

Software for Design, Optimization and Analysis of Optical Systems, Thin Films and Illumination Systems

# **Reference Manual**

Version 12.10



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# **Starting and Exiting OpTaliX**

OpTaliX can only be started from within Microsoft Windows. Within Windows, OpTaliX can be run by clicking on the OpTaliX menu item in the Program Group, double clicking on the OpTaliX desktop shortcut icon, double clicking on a lens file in Windows Explorer, or it can be run from a DOS prompt within a DOS window.

## 1.1 Starting OpTaliX from the Program Group

To start OpTaliX in Windows XP/Win7/Win10, click the **Start** button, click **Programs**, click the OpTaliX program group, and then click the OpTaliX menu item, as shown in Figure 1.1.



Figure 1.1: OpTaliX program group menu.

The OpTaliX program group also includes menu items for HTML-Help, Reference Manual, Tutorial and uninstalling OpTaliX. Note that two menu items for OpTaliX are found: **OpTaliX-Pro** and **OpTaliX-Pro-I**. Both versions, OpTaliX-Pro and OpTaliX-Pro-I, are functionally identical, except for the style of the windows.

# 1.2 Starting OpTaliX from Windows Explorer

The OpTaliX file format has been registered in Windows during program installation. This allows you to launch OpTaliX with a specific lens, by double clicking on the file (extension .otx) in Windows Explorer.

# **1.3 Starting OpTaliX from a DOS Window**

Open a DOS Window by clicking on the MS-DOS prompt menu item in the Program Group accessed by using **Start** - > **Programs**. From the DOS prompt on a 64-bit operating system, start OpTaliX by typing

C:> c:\Program Files\optalix-pro\optalix64p mylens.otx

respectively, if you have a network license, enter

```
C:> c:\Program Files\optalix-pro\optalix64pn mylens.otx
```

If OpTaliX was installed in a different directory than c:\Program Files\optalix-pro, the path to the OpTaliX executable must be modified accordingly. Specification of an OpTaliX lens file (mylens.otx) is optional. If omitted, OpTaliX starts with the recently used lens (i.e. the optical design which was in use during the last session). If specified, OpTaliX is launched and "mylens.otx" is automatically loaded.

# **1.4** Normal Exit from OpTaliX

- From the File menu, select Exit or click on the close window button  $\bowtie$  in the upper right corner of the OpTaliX main window.
- Select the main window (click on the title bar of the main window) and press the ESC-key.
- In the command line, type EXI or QUIT and press Return.

In all cases, you will be asked to confirm the exit. After you exit OpTaliX, you are returned to the operating system.

# 1.5 Forced Exit from OpTaliX

Normally an exit request invokes a dialog box asking to confirm exit. Immediate exit by bypassing the confirmation dialog box is accomplished from the command line or from a macro by

EXI Y

or

EXI Yes

The program is then terminated immediately.

# **Notational Conventions**

The following conventions are used throughout this manual:

- In syntax descriptions, [brackets] enclose optional items.
- In syntax descriptions, the vertical line | separates optional parameters within an option list.
- The apostrophe ' character encloses character strings which contain blanks. If there is no blank character contained in a string, the apostrophe may be omitted.
- OpTiX commands are emphasized by courier typeset.
- *ITALICS* refer to menue items of the GUI (graphical user interface)
- An ellipsis, "...", following an item indicates that more items of the same form may appear.
- The question mark "?" character, used within a command, activates additional dialog box information and/or settings.
- The semicolon ";" character separates command entries in the command line, i.e. it allows several command strings in a single line. A detailed description is given in the Macro section.
- The vertical bar "|" is not typed in any command, it means 'or' as in Yes | No, that is, you type Yes or No.
- The Dollar sign "\$" followed by a character denotes a short form of a directory path or part of it. These directories are created during installation.

\$i is the installation path, i.e. \$i may direct to c:\optalix or c:\programs\optalix
\$t is a temporary directory, e.g. c:\optalix\temp

\$c refers to the directory where coating files are stored, e.g. c:\optalix\coatings
\$g refers to the directory where glasses are stored, e.g. c:\optalix\glasses

• The asterix "\*" performs wildcard pattern matching in a given string.

# **Program Preferences**

Preferences are data associated with the program, not the lens. Change these settings only, if you know what you are doing. In particular, the directories must exist. Changes take effect immediately and it is not required to restart the program.

Preference settings are accessed from the main menu under File --> Preferences, or in the command line by entering "EDI PREF" (without the quotes). The settings are grouped into several categories, such as defining paths, behavior of the program (operations), windows, colours and other miscellaneous parameters.

## 3.1 Paths

The path information entered in the preferences section is used as a reference where files are searched first. Fig. 3.1 shows the corresponding dialog box.

### **POV Render Engine:**

Paths	Operations   Wind	dows   Colours   Miscellaneous   f at program start:	
PO	V-Render Engine	Files (x86)\POV-Ray for Windows v3.6\bin\pvengine.exe	Browse
Us	er Glass Catalogues	C:\ProgramData\OpTalX\glasscat\	
Co	atings	C:\Program Files\OpTalX-LT\coatings\	
Te	mp Dir.	C:\ProgramData\OpTalX\temp\	
Ma	eros	C:\ProgramData\OpTalX\macro\	
Us	er defined graphics	C:\ProgramData\OpTalX\macro\	

Figure 3.1: Preferences: Program default path settings.

OpTaliX provides an interface to the POV-Ray (Persistence of Vision) renderer, which is used to create almost photorealistic images of the optical system. POV-Ray is a separate program, which must be downloaded from http://www.povray.org and must also be separately installed. Once installed, the path where the executable of POV-ray resides must be entered into the path field. Use the "browse" button in the preferences dialog to select the path.

### **User Glass Catalogues:**

Specifies the path to user defined glass catalogues. These are typically Zemax AGF-glass catalogues that were converted to comma separated files (\*.csv) that are compatible to OpTaliX and using the CONVAGF command tool described in sect. 13.4.

### **Coatings:**

This field has been already defined during the installation of OpTaliX. It contains all thin-film coating files.

### **Temp Dir:**

Defines the path to a working directory used by OpTaliX for storage of intermediate data and other purposes. All files in this directory are normally used during runtime of the program only, however, these files are not deleted after program termination.

#### Macros:

Defines the path to the directory containing the macro files. The default extension is \*.mac. If empty, the macros will be stored and loaded by default from the currently active directory (i.e. the directory of the current system).

### User defined graphics:

Defines the path to the directory containing the files for *user defined graphics* (UGR). The default extension is \*.ugr. If empty, *user defined graphics* (UGR) will be stored and loaded by default from the currently active directory (i.e. the directory of the current system).

## 3.2 **Operations**

The settings in the "operations" tab determine the behaviour of the program (Fig. 3.2).

### Save current design as default on exit:

When the program is terminated, the current system is automatically stored as the "default" system. It is restored into memory at the next program start. This preserves design data between subsequent sessions.

### Put text output window to foreground ... :

Each time new output is written to the text window it will be raised to the foreground if this option is checked. This is particularly useful if many windows are opened and are obscuring the text window and the output contained in it.

### Warn if glasses are obsolete:

Issues a warning message when obsolete glasses are entered. These are glasses, which are no longer produced by a designated glass manufacturer.

### Align ray fans horizontally:

Normally transverse ray aberration fans and OPD fans are plotted with the pupil coordinate vertical. It is also possible to plot the pupil coordinate horizontal by checking the appropriate box. Selecting this option is merely a matter of personal preference rather than providing more detailed information.

### Refer fan aberrations to the physical coordinates of the stop surface:

When plotting ray aberration fans and OPD fans, the pupil coordinates are referred to the entrance pupil by default, that is where the rays intercept at the (fictitious) entrance pupil. Check this box if you want the plot coordinates to be referred to the physical ray intercept coordinates on the stop surface.

## Adjust surface apertures automatically:

It is sometimes required to adjust surface apertures, for example when system parameters (fields, system aperture) have changed or when the optical layout has changed after optimization. Apertures can be set manually on all surfaces as required by the beams going through the optical system using the SET MHT command. This task can be performed automatically such that surface apertures are always large enough. The oversize factor determines how much larger the apertures are set. For example, a factor 1.05 will oversize the apertures by 5% in relation to the required apertures.

## Blank command lines are mirrored in Text Output Window:

If this check box is enabled, entering a blank (empty) line in one of the two command lines produces a blank line in the text output window. This way, the user input in a command line is mirrored in the text output window, which allows adding extra blank (empty) in the text output window. This option has no effect on the command history window. The default setting of this option is disabled, i.e. blank command lines have no effect on text output.

## Selected surfaces in surface editor are highlighted in lens layout plot:

Check this box to highlight surfaces in the lens layout plot according to the focus in the surface editor. That is, clicking into any row (=surface) in the surface editor will show the corresponding surface in the layout plot in a different colour (typically blue). This feature helps identifying surfaces in the surface editor.

## 3.3 Windows

### Save position and size of windows on exit:

As windows can be interactively changed in size, position and can be minimized or maximized, checking this button saves the current settings of all windows if the program is terminated. The window settings will be restored at the next run of the program.

### Put text window to foreground when new output is generated:

Optical analyses may generate additional numerical output respectively informational or warning messages in the text window. If this check box is enabled, the text window will be put to foreground to immediately alert the user about a conflicting situation or simply to have additional information readily visible (i.e. in the foreground without needing to click on a particular window).

### Close all open windows on restoring a new optical system:

Prior to restoring a new optical system all currently open windows are automatically closed.

## **3.4** Colours

### Graphics window background colour:

This is an option which suits the personal taste of an user. Setting the background colour of **all** graphics windows to a different colour that the default (white) may help to reduce contrast or to make faint colours (like yellow) more visible.

🚨 Progr	am Preferences		-		$\times$
Pre only effe	ferences are data that are associated with the progra v, if you know what you are doing. In particular, the d ct immediately, if not otherwise noted.	m, not the lens. Ch rectories must exist	iange thes t. Changes	e settings : take	
Paths	Operations   Windows   Colours   Miscellaneous				
ा रा रा ा रा रा र	Save current design as default on exit. Always show sufface editor on program start, Warn if glasses are obsolete Align Ray Fan curves horizontally Refer fan aberration plots to physical coordinates of refer to coordinates in the entrance pupil. Refer OPD to reference wavelength Overlay through-focus MTF for all fields Adjust sufface apertures automatically. © Overs © Overs	stop surface. Leav ze by factor:   ze by fixed value:	re unchect 1.000	ked to	
	Blank command lines are mirrored in text output win Echo command line input in text output window. Selected surfaces in surface editor are highlighted ii	dow. n lens layout plot.			
	Help Cancel	OK			

Figure 3.2: Preferences: Operations, determining the behaviour of the program.

## 3.5 Miscellaneous

## Spot marker size:

Adjusts the size of markers used in spot diagrams. Marker size is defined in plot units (in mm) referred to the size of a standard A4 paper. See also the SPMS command for temporarily changing spot marker size within a session.

### **Contour Style**

Chose between two styles how contour plots are rendered: "*lines only*" or "*lines + area fill*". Since we consider this option a matter of personal preference, it is found in the general preferences rather than adjustable for each plot individually.

# **File Locations**

During operation OpTaliX creates intermediate files which are stored in the following directories, specific to each operating system:

## 4.1 Windows XP

User specific data are stored under Windows XP at:

c:\Documents and Settings\All Users\Application Data\OpTaliX.

## 4.2 Windows Vista / Windows 7 / Windows 10 / Windows 11

User specific data are stored under Windows Vista<sup>TM</sup>, Windows  $7^{TM}$ , Windows  $10^{TM}$  and Windows  $11^{TM}$  at:

c:\ProgramData\OpTaliX

## 4.3 Description of user-specific Files

In each of the user directories, depending on the operating system, a basic installation of OpTaliX contains the following files:

default	Without extension, this files contains the prescription data of the
	optical system in use after $OpTaliX$ was terminated. Upon
	restarting $OpTaliX$ , this system is automatically reloaded. The
	file format is ASCII.
optix.cfg	OpTaliX configuration file (ASCII format). Stores user-defined
	preferences as described in sect. 32.1.
coatp.asc	Standard ASCII file storing private (user-defined) coating mate-
	rials. A detailed description of the coating file format is given in
	sect. 32.3.
osp_priv.dat	ASCII file storing private (user-defined) optical spectra (i.e. spec-
	tral weights for calculating image performance).

# Definitions

## 5.1 Sign Conventions

Conventions are important because they define the frame of reference used for the results. These conventions are applied uniformly throughout the OpTaliX package. It is also important to adhere to strict sign conventions for curvatures and thicknesses (separations), which are determined according to the following rules:

- The radius of curvature of a surface is positive if the center of curvature lies to the right of the surface, otherwise it is negative. This rule is independent on the direction of the light, i.e. if the light travels from left to right (the default condition) or if it travels from right to left (after reflection from a mirror).
- The thickness (separation) of two consecutive surfaces is positive if (in axial direction) the next surface lies to the right of the current surface. If it lies to the left, it is negative.
- In case of tilted and decentered surfaces, the sign conventions apply to the local coordinate system of the current surface.
- A positive tilt means a rotation in counter-clockwise direction, a negative tilt is in clockwise direction.

## 5.2 Coordinate System(s)

The coordinate system used in OpTaliX is a left-handed system, with the Z-axis being the optical axis in most cases as shown in Fig. 5.1. The vertex of each surface is assumed to lie exactly on the Z-axis. The separation from one surface to the next is along the Z-axis.

## 5.2.1 Global Coordinate System

The global coordinate system is always located at the vertex of surface 1. Decenter/tilts applied to surface 1 do not change the global coordinate system. Fig. 5.2 illustrates this condition.

## 5.2.2 Object Coordinate System

The object coordinate system is a derived coordinate system of the global coordinate system. Object points ("fields"), for example, are always referred to the coordinate system defined by the object



Figure 5.1: Left-handed coordinate system used in OpTaliX

surface. In this way, the position and orientation of objects can be altered by changing position and orientation of the object surface (use XDE, YDE, ZDE, ADE, BDE, CDE commands applied to surface 0).

Using the object coordinate system may also be useful in defining extended sources (as opposed to point-like sources) in illumination calculations.

Note that the object coordinate system may be considered like the *local* coordinate system of any arbitrary surface. It is explained here to emphasize the its meaning for defining illumination sources.

## 5.2.3 Tilt Angles

The tilt angles in a tilted coordinate system are always given in degree. The sign of the tilt angles follows mathematical convention, i.e. it is positive for counter-clockwise rotation and negative for clockwise rotation. An Euler angle system is used in which each of the three tilt angles  $\alpha$ ,  $\beta$ ,  $\gamma$  takes place in the tilted coordinate system of the preceding tilt. Thus, tilting is non-commutative and undoing tilts must be applied in the reverse order.

Tilts and decenters are always applied to the local coordinate system of a surface.

## 5.3 Paraxial Conventions

The term paraxial means "near the axis". In this region, the linearized version of Snells' law is used:

$$n' \cdot u' = n \cdot u \tag{5.1}$$

with n = index of refraction and u = angle to the optical axis in radians. The computation of the paraxial entities (e.g. focal length, magnification, etc.) is performed using the ABCD matrix, which is defined as (see also Fig. 5.5):

$$\begin{pmatrix} n'u'\\h' \end{pmatrix} = \begin{bmatrix} A & B\\ C & D \end{bmatrix} \cdot \begin{pmatrix} nu\\h \end{pmatrix}$$
(5.2)

There are a few optical components (e.g. gradient index lenses, generalized aspheres) which are not well described by first order theory respectively very complex equations would result. In these cases, OpTaliX uses "parabasal" rays. These are real rays with very small angles to the optical axis (or the reference ray). The definition of the paraxial entities is given in Fig. 5.5.



Figure 5.2: The global coordinate system is always referred to the vertex of surface 1. If decenter and/or tilts are applied to surface 1, they are ignored (see right part of this figure).

## 5.4 Ray Coordinates

Rays are described by unit vectors with a starting point (X,Y,Z) and direction coordinates (CX,CY,CZ). The incidence angle *i* is always referred to the local surface normal at the ray intersection point.



Figure 5.3: Object coordinate system with reference to the global coordinate system.



Figure 5.4: Tilt angles and sign conventions for rotations about x-, y- and z-axis.







Figure 5.6: Definition of rays.

# **The Command Line**

## 6.1 General

OpTaliX has two modes of operation, either from the menu bar in the main window or from the command line. Although the menu provides an easy to use and easy to learn interface, the command line, which is found underneath the menu bar and in the text (output) window, offers a wider range of options and greater flexibility. All parameters and actions are accessible from the command line.

The syntax of the command line is universal throughout the program, since it is used for program control, for definition of optimization constraints and also in the macro language.

By default commands entered in the command line are reflected in the history window. Commands can also be "echoed" in the text window, if enabled by the "ECHO Y" command.

Any number of commands may appear in the command line, separated by semicolons ";". For example, two simple commands, which list the system data and plot a ray aberration fan, are:

lis fan

or, written in a single command line, separated by semicolons ";"

lis ; fan

## 6.2 Command Syntax

To a maximum possible extent, the command syntax used in OpTaliX is compatible with CODE-V commands. In addition, there are a few commands not found in CODE-V which describe dedicated OpTaliX features.

### 6.2.1 Qualifiers

Many of the commands accept parameters for surfaces, field, wavelength, zoom positions, rays, coefficients, pupils, sources, etc. The generic syntax is :
sk sijSurface (sk) or surface range (surfaces i to j),
also defines light source number. Distinction between surface number and lig
source number is made within command context.
fk   fi j Field (fk) or field range (field numbers i to j)
wk   wij Wavelength (wk) or wavelength range (color numbers i to j)
zk   zij Zoom position (zk) or zoom range (zoom position i to j)
$alt   ai \rightarrow Coefficient (alt) or coefficients range (range) it is used for holograms (HOE)$

- ck | ci. j Coefficient (ck) or coefficients range (range i to j, used for holograms (HOE), user-defined surfaces (UDC), and user-defined gradients (UDG).)
- pk|pi..jPupil number (pk) or range of pupils (= surface aperture) i to j
- lk | li..j Coating Layer (lk) or range of layers i to j
- gi Global reference surface number i

Thus, surface number, wavelength number, field number, zoom number, pupil number, coating layer, etc. must be preceded by its proper qualifier without spaces (e.g.  $\pm$  for surface,  $\pm$  for wavelength,  $\pm$  for field,  $\pm$  for zoom, etc.). A range of either surfaces, fields, wavelengths, rays, coefficients or pupils is specified by two consecutive dots "..."

If a range is specified on either surface, field, wavelength, zoom position, etc., the parameters are applied to all command items within the given range, e.g.

rdy s13 10.0	! sets radii of surfaces 1 to 3 to 10.0
yan f24 2.5	! sets Y-angle of fields 2 to 4 to 2.5 (degree)
spd f3 w2 z34	! analyzes the (RMS) spot diameter at field 3, wavelength number 2
	and zoom positions 3 to 4.
y s7 f1 w1 g2 0 1	! Outputs Y coordinate of a ray at surface 7, field 1, wavelength 1, in
	global coordinates referred to local coordinate system of surface 2

#### 6.2.2 Special Surface Qualifiers

There are special surface qualifiers for object surface, stop surface, image surface and *all* surfaces, which may be specified as

sofor object surface,ssfor stop surface,sifor image surface,saall surfaces.

The following commands are synonymous:

thi	sO	100	thi	SO	100							
cir	s5	12	cir	SS	12	!	assuming	surface	5	is	the	stop.
rdy	s8	-300	rdy	si	-300	!	assuming	surface	8	is	the	image.

#### 6.2.3 Variable Qualifiers

Qualifiers for surface, field, wavelength or zoom position may also be combined with variables. For example, thickness on surface s2 may also be defined by

\$x = 2 thi s\$x ... This feature may be understood as concatenating "s" (without the quotes) and the value of x. With the example given above,

s\$x is interpreted as s2 f\$x is interpreted as f2 w\$x is interpreted as w2 z\$x is interpreted as z2

These constructs are available in commands, macros and within lens database items (LDI).

#### 6.2.4 Entering and Changing Data

Entering and changing data is accomplished by a free format command syntax which is similar to CODE-V commands in many (but not all) respects. The main features of the command syntax are:

- It is uniform throughout OpTaliX and to a maximum possible extent compatible to CODE-V,
- it is flexible to support future needs,
- it uniformly uses blanks as delimiters,
- the command parameters can be used in any sequence,
- commands can be annotated by semicolon (;) separator.

All commands are case insensitive, i.e. the commands

RDY S1 34.5 rdy s1 34.5 Rdy S1 34.5

are interpreted in the same manner. All parameters are separated at least by one blank. Multiple blanks are treated as a single blank, i.e. the commands

RDY S1 34.5 rdy S1 34.5

are identical.

# 6.3 Surface Pointer

As the name implies, a surface pointer directs to a designated surface in the optical system. Use of a surface pointer allows simplified entry of construction data (such as radii of curvatures, thicknesses, etc). The surface pointer is set by the command

sk

where k denotes a surface number. Thus, sk means you should type s4 or s17, where 4 or 17 is the desired surface number. The actual position of the surface pointer is indicated in the prescription listing (see LIS command) by the > character right to the surface number . For example, the commands

s3 lis

#### produce the output

# TYPE	RADIUS	DISTANCE	GLASS	INDEX	APE-Y	AP	CP	DP	ΤP	MP	GLB
1 S	31.9354	4.90200	LAK9	1.694019	17.00*	C	0	0	0	0	0
2 S	95.0214	0.22600		1.000000	16.36	С	0	0	0	0	0
3>S	18.9471	5.42100	LAK9	1.694019	13.38	С	0	0	0	0	0
4 S	51.7823	2.82700	SF8	1.694169	12.29	С	0	0	0	0	0
5 S	12.8019	6.84900		1.000000	8.58	С	0	0	0	0	0

In second and succeeding references to the same surface number the surface qualifier can now be omitted, if desired. For example,

s3 rdy 100 thi 5.2

#### is fully equivalent to

rdy s3 100 thi s3 5.2

That is, in absence of a surface qualifier, the surface specified by a previous sk command is used. Note that the surface pointer is set to surface 1 on restoring a new optical system.

The current setting of the surface pointer can be queried by the command

s?

# 6.4 Surface Qualifiers and Arithmetic Expressions

Surface qualifiers (NOT field, wavelength, zoom or pupil qualifiers) also accept arithmetic operators, "+", "-", "\*" and "/". This is particularly useful in conjunction with the special qualifiers so, ss and si but also works for regular surface qualifiers, like s3 or s16. The following examples indicate valid usage of arithmetic operations on surface qualifiers:

si-1	surface before the image surface,
ss+1	surface after the stop surface,
so+2	denotes the second surface (object surface = surface 0 plus two surfaces),
s3i-1	denotes a range from surface 3 to the surface before the image surface,
s2s+1	denotes a range from surface 2 to stop surface plus one surface.
ss-1s+1	denotes a range from the surface before the stop surface to the surface after
	the stop surface.
ss-1ss+1	same as above
s47-2	surfaces 4 to 5
s3s4*2	invokes multiplication on surfaces, resulting in surfaces 3 to 8.
s4/2i-2	invokes division, resulting in surfaces 2 to image surface less 2.
s3-2+4	multiple operators are permitted.
s3+sqrt(4)	functions may be used, here resulting in surface 5. Note that only integer
	value should be used. Float numbers (albeit permitted) may lead to unpre-
	dictable results due to rounding effects.

Invalid surface or surface range qualifiers:

ss+-2	operator follows operator.
s3.5	surface range requires two consecutive dots.

## 6.5 Functions and Arithmetic Expressions

Numbers entered in the command line can also be arithmetic expressions or functions. In this way, it acts like a pocket calculator. For example, the entries

rdy s1 100 rdy s1 2\*(40+20)-20 rdy s1 sqrt(10\*\*4)

are all equivalent. Note that blank characters are not allowed in arithmetic expressions, except where enclosed in brackets. Expressions may also be copied from the clipboard directly to the command line. The functions and operators recognized are shown in table 6.1:

Functions	Operators
COS	+
sin	_
tan	*
exp	/
log	**
log10	^
logn	
sqrt	
acos	
asin	
atan	
cosh	
sinh	
tanh	
besj0	
besj1	
besjn	
anint	
aint	
abs	

Table 6.1: Functions and operators recognized by OpTaliX. See also section 26.2

In the command line brackets and correct order of operation are also recognized. In trigonometric functions, the argument must always entered in radians and inverse trigonometric functions report angles in radians. For example to compute  $sin(30^\circ)$ , it must be entered as sin(30\*3.14159/180). This form can be simplified by defining constants or variables and using them in arithmetic expressions

```
#define rad 3.14159/180
sin(30*rad)
or
@rad == 3.14159/180
sin(30*@rad)
```

Further details are given in chapter 26 (Macro Language).

## 6.6 Lens Database Items

Lens database items (LDI) are specifications of values which may be retrieved from the current optical system. Virtually anything that can be entered in the command line has a corresponding lens database item (see also chapter 27). All references to lens database items must be enclosed in rectangular brackets [], even if there are no qualifiers. Within the brackets, the syntax for database items is identical to the syntax used for command line input.

Examples:

```
thi s2 [EPD] ! sets thickness s2 equal to entrance pupil diameter
cuy s3 -[cuy s4] ! curvature on surface 3 is equal to minus the
! curvature on surface 4
```

Database items can be combined with arithmetic operators to form an arithmetic expression anywhere a numeric data entry is expected.

```
fno [EFL]/[EPD] ! sets F-number
thi s3 2*sqrt(3)*[thi s1]
```

Note that pre-defined functions (sin, tan, sqrt,...) and specification of lens database item references are case insensitive. For example, the following expression given in upper case, lower case or mixed case are valid:

```
thi s3 2*sqrt(3)*[thi s1]
THI S3 2*SQRT(3)*[THI S1]
thi S3 2*SqrT(3)*[thi S1]
```

See also a detailed explanation of the macro capabilities in chapter 26 and the lens database reference in chapter 27.

# 6.7 The Question Mark Symbol (?)

Most of the commands accept the "question mark" symbol "?", which allows a dialog based modification of relevant parameter. For instance, the fan (rim ray) plot may be entered in two ways:

זא גריד		plots the fan (rim ray) aberrations without asking for a scaling parameter
FAN		(the default or previously applied scaling factor is used).
Fan ?	2	invokes a dialog box to edit the aberration scaling factor prior to plotting
	•	the fan aberrations.

## 6.8 Rules for Command Entry

- Always separate parts of OpTaliX instructions with one or more blank characters (blanks).
- Never put spaces between command words, qualifiers, ranges or numbers. For example, LIS or S3 are valid entries, L IS or S3 (with blanks enclosed) are not.
- Upper and lower case letters can be used. OpTaliX ignores cases such as THI = tHi = thi.
- Arithmetic expressions such as 2\*3+5 must not contain blanks, except where enclosed in parentheses (). For example, 2\*3+5 and (2\*3 + 5) are equivalent, whereas 2\*3 + 5, (without the parentheses) are interpreted as two separate expressions.
- No spaces are permitted within numerics.
- Numeric input is defined as follows: Integers or floating point values with or without leading sign (+,-) or leading zeros, such as +0.5, .5, 5E-1, -2D-10, etc. (see also section 26.2).
- Always precede a surface number, field number, zoom number, wavelength number, etc. with its corresponding qualifier prefix (S for surface, W for wavelength, Z for zoom position, etc.), without spaces. For example, S3, W5 are valid entries, S 3 (with blanks) is not. O, S and I (for object, stop and image) are valid surface numbers. Examples: SO, SI, SS. Addition, subtraction, multiplication and division can be used on surface qualifiers only as in SI-1, SS+4, s3\*2, etc.
- Never add additional characters to command or qualifier words. For example, LIS is correct, LIST is not.
- Strings containing spaces, semi-colons ";" or ampersands "!" must be enclosed in single or double quotes.
- Continuation of commands with the ampersand character "&" is only possible in macros. This feature is not available in the command line.
- Multiple commands within a command line must be separated by the semicolon character ";".

7

# **Configuration and System Data**

In the terminology used throughout the manual, *system or configuration data* are data that pertain to the whole lens or describe its conditions of use. For example, typical system/configuration data, among others, are aperture, field of view and wavelength. These are attached to the lens data and are saved with the surface data.

# 7.1 Setting up a new lens system

Setting up a new lens system from scratch means that the previous system is deleted from memory, all old lens data is destroyed. An "empty" system is created which contains only two surfaces, the object surface and the stop surface. Reasonable default values are initialized. The command LEN is not necessary prior to restoring a lens from the library. This is done internally by the program. Optical surfaces may be added appropriately by the INS-command.

LEN	Set up a new lens. Initializes all surface parameter and defaults for a new lens. All old lens data is destroyed.
DIM I/M	Dimensional System. $M =$ millimeter (default), $I =$ inch
RDM yes/no	Select radius or curvature mode. Use radii (yes) instead of curvature (no) as the basic shape representation of a surface (default = yes). This option only works in command mode. In the surface spreadsheet editor only radii are accepted.

# 7.2 Saving and Restoring Lens Data

PES [file spec]	Restore lens data from file_spec.
KES [IIIe-spec]	Example: res c:/optix/test.otx
	Save lens data in file_spec. The complete path (directory
	and file name) must be specified. If file_spec is omitted,
SAV [file spec]	the existing file will be overwritten.
SAV [IIIe_Spec]	Examples:
	sav c:/optix/test.otx
	sav ! overwrites existing file.
WRL file_spec	Save lens data in Code V sequential format. See also sect.
	30.1.

# 7.3 General Lens Data (Configuration Data)

General lens data (or configuration data) define the usage of an optical system. These include specifications on fields, wavelengths and aperture, as well as a few special data such as afocal switches or methods of ray aiming.

The commands for editing/defining system configuration data are:

EDI CNF, or	
EDI CFG	Edit Configuration Parameter. A dialog box is opened.
EDI FLD	Edit Field Parameter. A dialog box is opened.
EDI LAM	Edit Wavelength Parameter. A dialog box is opened.
EDI ZOO	Edit Zoom Parameter. A spreadsheet is opened.
AFO yes  no	Afocal switch. Specifies that this is an afocal system where the exiting beam is nominally parallel (image is at infinity). This model assumes that a perfect lens is placed after the last surface (although the user does not explicitly need to specify this ideal lens, this is automatically done internally). The focal length of the ideal lens is pre-set to 1000mm, i.e. an aberration of 1 mm is equivalent to 1 mrad in image space.
TIT 'string'	Enters a title (max. 256 characters). The title is displayed in the lens layout plots and the system prescription.
RDM yes no	Select radius or curvature mode. Use radii (yes) instead of cur- vature (no) as the basic shape representation of a surface. (de- fault = yes)
SET MAG mag_value	Set magnification. Changes the object distance required to sat- isfy <i>paraxial</i> magnification of mag_value. This is a static (one-time) adjustment. In order to adjust magnification perma- nently (dynamically as the system changes), use the RED solve (page 109).

#### 7.3.1 Fields / Object Points

In optical design, the term "fields" describes the entity of object points used for calculating the performance of an optical system. Thus, a "field", or field point, is just the location of an (infinitesimally small) object point defined at the object surface (respectively referred to the object coordinate system (page 29)). For reference see also the object coordinate system.

Another way to specifying objects is by defining extended emitting sources, which are mainly used in illumination analysis. See chapter 15, page 305 for a detailed treatment of this type of sources.

Resorting to **point** objects, the number of field points (objects) is unlimited. Initially, a maximum number of 30 field points is assumed, however, this value can always be increased to any arbitrary value using the MAXFLD command. Fields can be specified independently in X- and Y-direction in terms of object height (XOB, YOB), paraxial image height (XIM, YIM), real image height (XRI, YRI) or angles (XAN, YAN) in the object space. Fig. 7.1 shows the four types of defining fields.



YOB = -L \* tan(YAN)



EDI FLD	
	Invokes a dialog box to enter X-field, Y-field, field type,
	and number of field points. Command line input is given
	by the commands below.
NFLD num_fields_used	Number of field points in use for performance analysis.
	This command must not confused with MAXFLD (see
	below). Also note that you should set NFLD to the max-
	imum number of fields before saving the system, other-
	wise field data larger than num_fields_used will be
	lost.
MAXFLD max_fields	Maximum number of field points (objects). This com-
	mand does not affect the number of fields in use for per-
	formance analysis (see NFLD command), it merely sets
	the maximum number of <i>allocated</i> fields.
XAN [fij] x_angle1	
x_angle2 x_angle_n	Field angle (in degree) in X-direction, referred to Z-
	Axis. The number of entered field angles also sets the
	number of fields during performance analysis.
YAN [fij] y_angle1	
y_angle2 y_angle_n	Field angle (in degree) in Y-direction, referred to Z-
	Axis. The number of entered field angles also sets the
	number of fields during performance analysis.
XOB [fij] x_obj1 x_obj2	
x_obj_n	Object coordinates (X) for finite object distances. The
	number of entered field angles also sets the number of
	fields during performance analysis. <b>XOB data will be</b>
	interpreted as X-field angles if the object is at infinity.
	See also notes below.
	continued on next page

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YOB [fij] y_obj1 y_obj2 y_obj_n	Object coordinates (Y) for finite object distances. The number of entered field angles also sets the number of fields during performance analysis. <b>YOB data will be</b> <b>interpreted as Y-field angles if the object is at infinity.</b> See also notes below.
<pre>XIM [fij] x_image1 x_image2 x_image_n</pre>	Image coordinates (X), defined in the <i>paraxial</i> domain. The number of entered fields also sets the number of fields during performance analysis.
YIM [fij] y_image1 y_image2 y_image_n	Image coordinates (Y), defined in the <i>paraxial</i> domain. The number of entered fields also sets the number of fields during performance analysis.
XRI fij x_real_img_ht	Compute X-object height based on real image height. Object heights are continuously adjusted as the lens changes. Ensures that the real chief rays (at the refer- ence wavelength) hit the image surface at the specified image heights. Not applicable in afocal (AFO Y) sys- tems.
YRI fij y_real_img_ht n	Compute Y-object height based on real image height. Object heights are continuously adjusted as the lens changes. Ensures that the real chief rays (at the refer- ence wavelength) hit the image surface at the specified image heights. Not applicable in afocal (AFO Y) sys- tems.
FTYP field_type	<ul> <li>Field type. This is a complementary command to change the field type specification (i.e. XAN, YAN, XOB,YOB, XIM,YIM).</li> <li>Field type is defined as : <ol> <li>= specifies angles (XAN,YAN)</li> <li>= specifies object coordinates (XOB,YOB)</li> <li>= specifies paraxial image coordinates (XIM,YIM)</li> <li>= specifies real image coordinates (XRI,YRI).</li> </ol> </li> </ul>
<pre>FWGT [fij] fweight1 fweight2 or WTF [fij] fweight1 fweight2</pre>	Field weight, an integer value between 0 and 100.
FACT [fij] 0/1	Field activation. A particular field point may be excluded from analysis, i.e. it is not active. 0 = inactive, 1 = active.
	continued on next page

continued from previous page	
CLS FLD [fk fij] [colourn]	Selects the colour list used for fields in graph- ical output (e.g. VIE). Input of fewer colours than the number of fields uses the last colour entered for the rest of the fields. With no colours specified, colours are set to default settings. Examples: cls fld red gre blu ! defines red, green and blue for the first three fields. cls fld ! no colours specified, default field colours are selected. cls fld f3 red ! change plot colour for
	See also names of predefined colours and their definition in sect. 28.1, page 489.

#### Notes:

- For objects at infinity (i.e. object distance is  $\geq 10^{20}$ ), object coordinates (either entered by XOB,YOB commands or defined by 'FTYP 2' command) are specially handled. Field values are then interpreted as field *angles* instead of real object coordinates. It is obvious that object coordinates must also be very large for infinitely distant objects (i.e. THI  $\leq 0$  is  $\geq 1.E20$ ). For example, an apparent field angle of  $30^{\circ}$  would require an object height (OBY) of  $tan(30) * 10^{20} = 5.77E19$ . This may lead to a loss of internal computational accuracy and the program therefore interprets field values for infinitely distant objects as field *angles* (in degree).
- Field specifications can be entered in any order. It is not required that they be ascending or descending values.
- If the system is rotationally symmetric, only Y-field specifications should be used, i.e. X-field components are zero. The program checks for symmetry condition about the Y-axis to reduce computing time.
- Object space field specification (XOB/YOB or XAN/YAN) are recommended for systems with decentered surfaces.
- Paraxial image space field specification (XIM/YIM) is useful for zoom systems with constant image size across zoom positions. This eliminates the need to zoom field specifications.
- Real image space field specification (XRI/YRI) is useful when exact image points are desired. Includes effects of distortion, which is particularly useful in zoom systems where distortion can vary across zoom position.

#### 7.3.2 Astigmatic Objects

Simulates an astigmatic shift in the emitted light which some sources, such as laser diodes, have. This option is only available for finite object conjugates.

ASF delta_f_microns	Astigmatic focus shift in microns. Shift of sagittal source (i.e. X/Z-plane) from the tangential source (Y/Z-plane). If 0 is entered for ASF, the astigmatic shift is disabled. The astigmatic focus is always defined in microns and is always measured along the chief ray.
ASO angle_degree	Orientation (in degrees) of astigmatic focus shift. 0 corresponds to shifted source oriented with X-axis.

In gain guided laser diodes, light appears to diverge from different points, depending on the orientation considered. Light perpendicular to the active layer emits from the front face of the diode, whereas light in the plane of the active layer is emitted from a virtual point located between  $20\mu m$  to  $30\mu m$ behind the emitting window (in negative Z-direction).



Figure 7.2: Geometry of astigmatic focus shift in a laser diode.

#### 7.3.3 Wavelength Definition

The number of wavelength is limited to 11. The order and sequence of the wavelengths may be arbitrary. There is always one specific wavelength which serves as reference wavelength. It is used to define first order (paraxial) properties, pupil definition, image plane location, etc.

EDI LAM	Invokes a dialog box to enter wavelength, weights, number of wavelength and reference wavelength. The dialog box is shown in Fig. 7.3
	shown in Fig. 7.3.
	continued on next page

continued from previous page	
WL lam1 lam2 lam3 lam11	Wavelength definition. Enter up to 11 wavelengths (in $\mu m$ ) in any order. The number of entered wavelength values also sets the number of wavelength during performance analy- sis. Example: w1 0.546 0.48 0.7 sets 3 wavelength (colours).
NWL no_of_wavelengths	Sets the number of wavelengths used in the system.
REF ref_w	Sets the reference wavelength. It designates which of the WL wavelengths is to serve as the reference wavelength for all first order properties and monochromatic aberrations. Example: REF 2
WTW weight	<ul> <li>Weights for corresponding wavelengths. (Specifies relative spectral intensities). The values given are integer numbers and range from 0 to 100.</li> <li>Example: WTW 50 100 75</li> <li>Note: the wavelength weights may also be edited in a dialog box using the command EDI LAM (see above).</li> </ul>

#### 7.3.4 Optical Spectrum

Rather than enter wavelength/weight pairs explicitly you can store wavelength data as an *optical spectrum*. An optical spectrum is the collection of wavelengths, weights, and reference wavelength stored with a user-definable name for later retrieval. This feature is particularly useful in zoom/multi-configuration systems utilizing different spectral channels. Different optical spectra (i.e. wavelength/weight combinations) may be assigned to each zoom position in a single command.

OSP spectrum_name [?]	Loads a predefined optical spectrum and automatically sets wavelengths, corresponding wavelength weights and refer- ence wavelength. The number of wavelength to be used must be previously set by the NWL command (see above). A list of available optical spectra is given below. Examples: osp photopic ! selects visible (daylight, photopic) spectrum. osp ? ! invokes a dialog box to interactively set the optical spectrum (see Fig. 7.3).
OSP PLANCK temp_degK	Sets the optical spectrum according to the spectral radiance of a black body using Planck's law. A third parameter, the temperature of the black body in Kelvin is expected. This command uses the currently defined wavelengths and only sets wavelength weights! This option is currently only available from the command line. Example: osp planck 6000 ! Sets wavelength weights ac- cording to a black body spectrum at 6000K.
	continued on next page

continued from previous page	
SAV OSP spectrum_name	Save optical spectrum (wavelengths, weights and refer- ence wavelength) under spectrum_name. Use OSP command to assign a saved spectrum to the system con- figuration data.

#### List of predefined optical spectra:

Spectrum name	Description
<b>'</b> an	Spectral sensitivity of a typical panchromatic film.
Photopic	Relative sensitivity of the human eye for daylight illumination (photopic
	vision).
Scotopic	Relative sensitivity of the human eye under conditions of dark adapta-
	tion (scotopic vision)
MWIR	Medium wave infrared, $3\mu m$ - $5\mu m$ waveband
/LAM	Same as "Photopic"
Pan Photopic Scotopic MWIR VLAM	Spectral sensitivity of a typical panchromatic film. Relative sensitivity of the human eye for daylight illumination (photopic vision). Relative sensitivity of the human eye under conditions of dark adaptation (scotopic vision) Medium wave infrared, $3\mu m - 5\mu m$ waveband Same as "Photopic"

#### Dialog based editing of optical spectra:

Wavelengths, weights and reference wavelength can also be edited in a dialog box which is accessed from the main menu *Edit/Configuration* and then selecting the *wavelengths* tab (see Fig. 7.3). The ensemble of wavelengths and corresponding weights constitutes an "optical spectrum". It defines the wavelength range and also the relative spectral intensities (weights) within that range. Weights are given by integer numbers, preferably between 0 and 100, but any other positive number is also accepted.

A set of predefined optical spectra may also be directly selected from the combo box in the right part of the dialog. Choosing one of the predefined spectra avoids entering each wavelength/weight pair manually. Once an appropriate spectrum has been selected, pressing the "Set" button underneath the graphical display of the spectrum will automatically set wavelengths, weights and reference wavelength.

#### Freeze optical spectrum:

When an optical spectrum is selected and applied to the system configuration, all wavelengths will normally be equidistantly scaled within the spectrum limits. If you wish to apply wavelengths exactly as defined and stored, check the "Freeze optical spectrum" check box in the wavelengths tab.

#### 7.3.5 System Aperture

The system aperture defines the aperture used for the whole lens. This definition must not be confused with surface apertures (see 8.33 on page 167).

The system aperture may be defined in various ways, for example by

- NA, the numerical aperture in the image space,
- NAO, the numerical aperture in the object space,
- EPD, the entrance pupil diameter,
- FNO, the F-number,
- or by the physical stop semi-diameter.

Optical	System Config	uration		
Aperture	Fields Wav	elengths	General Asti	gmatic Object   Illum.Source
No.	of Wavelengths	5	•	Select Optical Spectrum (OSP)
	Wavelength	Weight	REF	
1	0.475000	15	C 1	
2	0.512500	44	C 2	
3	0.550000	102	€ 3	
4	0.587500	72	C 4	
5	0.625000	34	C 5	
6	0.000000	0	C 6	0.50
7	0.000000	0	C 7	
8	0.000000	0	C 8	MAM
9	0.000000	0	C 9	
10	0.000000	0	C 10	Freeze optical spectrum
11	0.000000	0	C 11	C. Set Save as Delete
			Spec	cific Help Cancel OK

Figure 7.3: Wavelength and optical spectrum editing.





Figure 7.4: Defining system apertures.

#### **Commands:**

FNO [zij zk] F_number	Define aperture by F-number in the image space. The stop diameter is adjusted to satisfy the F-number when the lens is changed. Note: The F-number is calculated by definition at magnification = $0$ (object at infinity).
DEL FNO	Delete previous F-number setting, so the stop diameter is no longer automatically adjusted.
	continued on next page

continued from previous page	
EPD [zij zk] entrance_pupil_diam	Entrance Pupil Diameter (EPD). This command sets the stop surface aperture dimensions to satisfy the entrance_pupil_diam condition. In case of a rectangular aperture, the EPD is defined as the diagonal of the rectangle, i.e. the surrounding circle. In case of an elliptical aperture, the EPD is the maximum value of the ellipse axes.
DEL EPD	Delete previous EPD (entrance pupil diameter) setting, so there is no subsequent adjustment of the stop diameter.
NA [zij zk] num_aperture_image	Define aperture by numerical aperture in the image space (at working magnification). It adjusts the stop diameter to satisfy the num_aperture_image requirement when the lens is changed.
DEL NA	Delete previous numerical aperture setting, so there is no sub- sequent stop diameter adjustment.
NAO [zij zk] num_aperture_object	Define aperture by numerical aperture in the object space (at working magnification). It adjusts the stop diameter to satisfy the num_aperture_object requirement when the lens is changed.
DEL NAO	Delete previous numerical aperture setting (in object space)
POF oversize_factor	Increases the dimension of the system aperture by a factor oversize_factor for the ray grid. The default factor is 1. POF only needs to be modified in systems showing significant pupil distortion, for example in wide-angle retrofocus systems.
	Related Command
NRD num_rays_diam	Number of rays across pupil diameter. Defines the size of the (rectangular) ray grid in the entrance pupil. NRD is ad- justable in $2^n$ steps, i.e. the ray grid may have sizes of $4^2$ , $8^2$ , $16^2$ , $32^2$ , $64^2$ , $128^2$ , $256^2$ , $512^2$ and $1024^2$ . The higher num_rays_diam is, the more accurate the results will be. However, the computing time will increase quadratically with increasing num_rays_diam. Although $1024^2$ rays are ac- cepted by the program, practical memory limitations make this option unlikely. Practice has shown, that grid sizes of $64^2$ or $128^2$ rays are very rarely required and $32 \times 32$ rays (the default in $OpTaliX$ ) are the best compromise between accuracy and speed. The ray grid is used in geometrical and diffraction anal- ysis, e.g. spot, wavefront, PSF, MTF, etc.

**Note:** The aperture definitions (NA, NAO, EPD, FNO) permanently adjust the stop diameter when system parameters change, unless aperture adjustment is deactivated by any of the commands DEL NA, DEL NAO, DEL EPD or DEL FNO. The stop aperture then remains fixed.

In case of non-circular *system* apertures, i.e. rectangular, elliptical or polygon system apertures, specifications of NA, NAO, FNO or EPD are always defined by the surrounding circle of the non-circular system aperture. This convention is illustrated in Fig. 7.5 on the examples of rectangular and polygon system apertures.



Figure 7.5: Definition of *system* aperture (not surface aperture!). Similarly, this also applies to elliptical apertures. NA, NAO, FNO and EPD are always referred to the surrounding circle of the complex system aperture shape.

#### 7.3.6 Pupil Apodization

Gaussian intensity distribution across the entrance pupil. In most cases, this feature is required to simulate a laser beam which is clipped at a certain level at the paraxial entrance aperture.

PUI intensity	Apodization of intensity across the (paraxial) entrance pupil
	with a gaussian distribution. intensity defines the intensity
	at the relative pupil coordinates of PUX, PUY. The peak inten-
	sity is 1 at the aperture center (PUX=PUY=0). The default is
	PUI 1.0 which corresponds to a flat (unapodized) intensity
	distribution.
PUX rel_ape_radius_X	Relative X pupil coordinate (normalized to the entrance pupil
	radius) at which the PUI value is reached. The default is PUX
	1.0
PUY rel_ape_radius_Y	Relative Y pupil coordinate (normalized to the entrance pupil
	radius) at which the PUI value is reached. The default is PUY
	1.0

An elliptical intensity distribution may be defined with different values for PUX and PUY. A gaussian intensity apodization, defined by the commands PUI, PUX, PUY, is evaluated by:

$$I(x_p, y_p) = e^{(\ln \text{PUI}) \left[ \left(\frac{x_p}{X}\right)^2 + \left(\frac{y_p}{Y}\right)^2 \right]}$$
(7.1)

with

 $I(x_p, y_p)$ Intensity $x_p, y_p$ entrance pupil coordinateXPUX \* (entrance pupil radius)YPUY \* (entrance pupil radius)

Eq. 7.1 normalizes the Gaussian apodization to 1 at the center  $(x_p = y_p = 0)$  and at the value of PUI at the elliptical contour defined by PUX, PUY. Equal values for PUX and PUY designate a circular

apodization. PUX and PUY may have any value, except 0.

#### **Examples:**

A circular gaussian intensity distribution, with intensity 0.135 at the rim of the entrance pupil, is specified as

PUI 0.135 PUX 1. PUY 1.

An elliptical gaussian intensity distribution, with intensity 0.5 at relative pupil coordinates X = 1, Y = 0.7 is specified as

PUI 0.5 PUX 1. PUY 0.7

#### Notes on entrance pupil apodization:

- Entrance pupil apodization should be regarded as a property of the incoming beam rather than the lens.
- Apodizing that occurs at surfaces inside the lens should be represented by 'surface intensity filters' stored in INT-files as described in section 8.28.5.
- Entrance pupil (and surface-based INT) apodization is included in all geometrical and diffraction analysis options.
- PUX, PUY are defined on a plane perpendicular to the chief ray at a given field. For an on-axis object point, the apodizing plane is also perpendicular to the optical axis, however, for off-axis field points the apodizing plane tilts in the same direction and by the same amount as the corresponding chief ray for that field.

#### 7.3.7 Defocus

	Defocus value. The defocus defines the offset of the physical image plane from the paraxial focus. A negative value of DEF means that
	the physical focus is intrafocal (left) from the paraxial focus, and vice
	versa.
	Defocus is only taken into account for "PIM yes". If paraxial
DEF defocus	image solve is turned off (PIM no), DEF (defocus) has no effect.
THI si defocus	The distance to the paraxial image, however, is still displayed for
	<b>information only!</b> See also Figs. 7.6 and 7.7 for a representation of
	DEF and the associated data BFL and IMD.
	Note that the defocus may also be defined as the distance on the im- age surface (THI si). That way, DEF and THI si are identical.

Typically 'defocus' is used to account for (spherical) aberrations in an optical system for finding the optimum focus. As shown in Fig. 7.6 below, the lens exhibits significant amount of spherical aberration. Selecting the exact paraxial image plane apparently does not yield the optimum focus for



Figure 7.6: Representation of 'defocus' with respect to paraxial image. Defocus (DEF) is always measured from the *paraxial* image to the *physical* image surface at used conjugation. The image distance (IMD) is always measured from the last surface to the physical image surface.

which aberrations are minimized. Introducing an appropriate defocus term moves the *physical* image surface away from the paraxial image surface to the location of minimum circle of confusion.

Image distance (IMD) and defocus (DEF = THI si) are displayed in the surface editor (invoked by EDI SUR) as shown in Fig. 7.7. The defocus value can only be modified if "PIM Y" is set, otherwise (PIM N) defocus settings have no effect.



Figure 7.7: Display of image distance (IMD) and defocus (DEF) in the surface editor.

REM	The REM command allows entry of up to 4 lines of text which are stored with the lens system. The comments are
	displayed with the system data listing and with the lens
	cross sectional view.
TIT 'string'	A title of the lens system, enclosed in apostrophes, can be
	entered. Up to 256 characters are allowed for 'string'.
COM sij comment_string	Enter a descriptive text (up to 80 characters) per surface(s)
	sij.
SLB sij comment_string	As above, enter a descriptive text (comment) containing up
	to 80 characters per surface(s) sij. This command is
	equivalent to the COM command, but has been added for
	Code V compatibility.

### 7.3.8 Remarks and Comments

# 7.4 Ray Aiming Methods

Ray aiming is the method of determining start coordinates for selected fields. Ray aiming can be controlled by three parameters, RAIM, RAIT and RAIS. The RAIO command is obsolete (though still available) but use is discouraged. In general, the default settings for these three parameters need not be altered, but may accelerate ray generation in a few special cases.

	Ray aiming modes:				
	ENP Rays are aimed at the paraxial entrance pupil.				
	STO Rays are aimed to the physical stop surface.				
	This is the default mode.				
	TEL Telecentric ray aiming.				
RAIM [	OMN Omni-directional, i.e. rays are launched from				
ENPISIO ILLIOMN ]	a point source into arbitrary directions within				
	$4\pi$ directional space. See also the commands				
	OMN MIN and OMN MAX below.				
	A detailed description on ray aiming methods is given below.				
RAIT tolerance					
	Ray aiming tolerance. Only applicable for RAIM STO. The				
	default ray aiming tolerance is 0.001 and is understood as a				
	fraction of the aperture radius. For example, RAIT 0.001 on a				
	5mm aperture terminates ray iteration if the error on the desired				
	ray coordinate is $< 0.001 \cdot 5mm$ , i.e. $< 0.005mm$ .				
RAIS max_search_step					
	Ray aiming maximum step. Limits the step size during iteration				
	for finding the start coordinates of a ray. max_search_step				
	is defined in fractions of the entrance aperture, i.e. 1.0 cor-				
	responds to a step equal to the entrance pupil radius. Smaller				
	values improve the probability of successful ray finding, in par-				
	ticular for systems with large pupil aberrations (for example				
	wide-angle systems), however, speed of convergence may be				
	reduced. Larger values accelerate ray iteration speed but ray				
	aiming may fail on unusual systems. Reduce RAIS in such				
	cases. The default value of RAIS is 5.				
	continued on next page				

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RAIO 0 1	Ray aiming option, now obsolete (but still available). RAIO 1 is equivalent to RAIS 0.2. This allows switching between normal ray aiming mode (RAIO 0) and a more accurate (but signifi- cantly slower) mode (RAIO 1). The default setting is RAIO 0. The mode RAIO 1 should <b>only</b> be enabled if the 'normal' ray iteration mode fails, which is <i>very</i> rarely the case. RAIO 1 does a finer search and also checks for false convergence conditions. For example, in some wide-angle systems, it may be advisable to switch to RAIO 1. Use this switch with care! This setting is saved with the prescription data.
OMN MIN MAX angle_deg	Specifies minimum (MIN) and maximum (MAX) angles in de- grees at which rays can be launched in the omni-directional ray aiming mode. Requires that RAIM OMN is set, otherwise this command has no effect.
	Examples: OMN MIN -80 ! minimum omni-directional angle is -80° OMN MAX 130 ! maximum omni-directional angle is 130°
EPX Y N	Ray aiming could fail when decentered or tilted surfaces in front of the stop surface could distort the entrance pupil. The EPX command supports the ray iteration convergence by first doing an inverse ray trace from the stop to the outside world, so that better start coordinates for the iteration can be found.
	EPX Y ! pupil distortion is considered in ray iteration EPX N ! pupil distortion is ignored.
	In case of decentered or tilted surfaces in front of the stop, there is no iteration advantage and it is recommended to turn this option off (EPX N).

The ray aiming mode determines the generation of the start rays in the object space. By default, ray aiming is performed for all wavelengths in use. Because ray aiming for all wavelengths is time consuming, an option to confine ray aiming to the reference wavelength is given in the configuration dialog. Select *Edit - Configuration* from the main menu. In the *Aperture* tab, disable the check box "Ray aiming at ALL wavelengths". Ray aiming is then performed at the reference wavelength only.

Currently there are four modes available to define start rays from an object point towards the pupil of a system:

#### 7.4.1 ENP: Paraxial entrance pupil mode:

Rays are aimed to the *paraxial* entrance pupil. This mode does not account for pupil aberrations and is independent on tilted and decentered surfaces in the system. Since only paraxial quantities are used, it is the fasted mode. However, paraxial ray aiming may fail in systems with noticeable pupil aberrations, such as in wide angle systems or systems with large numerical aperture. If this occurs, use the STO ray aiming method described in the next section.

## 7.4.2 STO: Stop Surface Mode

Rays are aimed to the physical boundaries of the stop surface, independent of its shape (circular, elliptical, rectangular, etc.). This is an iterative process and therefore consumes more time. It also takes tilted and decentered surfaces and apertures into account, as well as vignetting caused by undersized surface apertures.

The effect of ray aiming mode "STO" is neatly observed with wide-angle lenses which exhibit strong pupil distortion. Fig.7.8 gives an example of this effect. If rays are aimed to the paraxial entrance pupil, i.e. RAIM ENP, they will not hit the real stop surface at all for some field angles. This is due to the fact that the axial position of the entrance pupil varies strongly with field angle. Since paraxial quantities do not account for field dependent effects, solely aiming to the *paraxial* entrance pupil will fail in most wide-angle systems.

Therefore, in using RAIM STO, the correct start coordinates of the rays are exactly traced in an iterative process, such that size and position of the stop are always exactly found.



Figure 7.8: Ray aiming methods. Rays aiming to the paraxial entrance pupil (RAIM ENP) will not hit the stop surface at the corresponding coordinates. RAIM STO takes account for pupil aberrations in centered and decentered systems by iterating for the exact start coordinates.

#### 7.4.3 TEL: Telecentric Mode

Systems having an infinitely distant entrance pupil are best modelled in the telecentric mode. The initial direction of chief rays in the object space is always parallel to the optical axis. The telecentric mode requires systems with a *finite* object distance and the angular subtense of the beam emerging the object must be defined by the numerical aperture (see NAO command).

Note, that telecentric beams do not necessarily go through the center of the stop. Since the stop surface is always limiting the beams (independent of the FHY setting on the stop surface), it may be likely that the stop surface truncates the beams in an unwanted manner. The aperture dimensions of the stop should be appropriately oversized if such effects are not wanted.

#### 7.4.4 OMN: Omni-directional Mode

In some systems it is necessary to launch rays into arbitrary directions, irrespective of stop position or definition of the system aperture (such as NA, EPD, FNO, etc). This can be a valuable option,

for example in condensor systems or illumination systems in which sources irradiate into the full  $4\pi$  angular space.

For example, Fig. 7.9 shows an elliptical reflector where rays are launched from a point object at angles greater than  $\pm 90^{\circ}$ , i.e. rays also exit the source in opposite direction to the positive Z-axis. This is normally not possible with the standard ray aiming (generation) methods ENP, STO, and TEL as described above.



Figure 7.9: Example of omni-directional ray aiming. See examples directory \examples\mirror\ellipsoid\_1.otx

The only parameters required for defining an omni-directional beam are the minimum and maximum angles (referred to the global coordinate system) at which rays can be launched from a point source. Fig. 7.10 illustrates an arbitrary condition. The allowable range of minimum and maximum source ray angles is from  $0^{\circ}$  to  $\pm 180^{\circ}$ .





In omni-directional mode, rays are generated such that their intersections with a sphere are equidistant, like with the degrees of longitude and latitude on the globe. This imposes some difficulties with some kinds of analysis plots. For example the results of ray intersection plots or illumination plots are always referred to the tangent plane at a given surface. Since it is impossible to convert a coordinate system based on spherical coordinates to a plane, distortion of a regular ray grid emitted from a point source is always distorted on a plane.

# 7.5 Afocal Systems

In an afocal system the principal points and focal points are at infinity, which does not imply that the object and image are at infinity. This condition requires special procedures to be used in ray tracing because tracing to infinity would create numerical problems. We will distinguish between afocal in the object space and afocal in the image space. While *afocal in the object space* is quite normal in many systems, *afocal in image space* is handled by *angular* ray aberrations instead of transverse ray aberrations in a finite image plane. To illustrate the concept of angular measures, we will consider a simple Fraunhofer-type telescope as shown in Fig. ...

A rim ray exits the system at an angle  $\alpha$  to the optical axis due to inherent aberrations in the system. Since the image is assumed at infinity (afocal in image space), the transverse aberration of the ray would also be infinity. At this point we will introduce the concept of a virtual "ideal" lens, which is placed at the exit of the system and helps us to convert the angular aberration of the ray to a finite measure. For simplicity, the focal length of the ideal lens is assumed 1000mm, thus converting an angle  $\alpha = 1mrad$  to a transverse aberration y' = 1mm.

The beauty of the "ideal lens" concept is, that we do not need to leave our world of transverse aberrations. If the system is afocal in image space, 1mm aberration in the focal plane of the assumed "ideal" lens corresponds to 1mrad angular ray deviation.

If the system is a focal (in image space), OpTaliX automatically does this conversion internally. It is not necessary to add an ideal lens after the optical system. The only command required to make a system afocal is

AFO yes

irrespective whether the focus is actually at infinity or not. All performance analyses (Spot, Fan, MTF, PSF, etc.) will then be given in angular aberrations (mrad) instead of transverse aberration (mm).

Optical path differences (OPD) will be referred to a plane wave in the exit pupil of the system. Since the focal length of the (internally used) ideal lens is always 1000mm, field sags are reported in diopters.

# 7.6 Vignetting

Vignetting in optical systems is defined by the shape and dimensions of the stop surface and by hard limiting (fixed) apertures on other surfaces using the FHY command. There can be as many fixed apertures as there are surfaces in the optical system. Fixed apertures are indicated in the system listing (see LIS command) by an asterisk (\*) character immediately following the aperture value.

SET VIG	Calculates vignetting factors VUX, VLX, VUY, VLY
	in accordance to the setting of fixed (hard limiting) sur-
	face apertures. Included for Code V compatibility. See
	also notes below.
DEL VIG [fij]	Delete vignetting factors for fields i to j.

For related commands, SET MHT and FHY see section 8.33.3 on page 171.

#### Notes on SET VIG Command:

Modelling of ray bundles in OpTaliX is solely based on hard-limiting (fixed) apertures on surfaces. Even though vignetting factors can be evaluated (SET VIG), they are reported for information only and do not have any impact on size and shape of light beams.

Since light beams are always calculated using real apertures, there is no risk of inconsistency and OpTaliX will always calculate the correct beam. In particular, rays shown in the lens layout plot actually represent the beam limits used for all performance analysis options.

A typical output of the SET VIG command is as follows:

VIGNETT	ING FACTORS:							
Field	VUX	VLX	VUY	VLY	UX	LX	UY	LY
1	-0.00011	-0.00011	-0.00011	-0.00011	6	6	6	6
2	-0.00002	-0.00002	-0.00003	-0.00010	6	6	6	6
3	0.00043	0.00043	0.17753	0.13093	6	6	11	1

Vignetting factors are given for each field separately. The UX, LX, UY, LY columns denote the surfaces which limit the beam. On the example given above, at field 3, surface 11 limits the upper Y-portion (UY) of the beam whereas surface 1 limits the lower Y-portion of the beam.

# **Surface Data**

8

Surface data include the typical lens prescription items such as radius of curvature, thickness (axial separation), glasses, etc. The numbering sequence starts with 0 for the object surface. The first surface of the optical system is surface 1 and, in a normal (sequential) system, the surface numbers increase monotonically in the order that rays strike them.



Figure 8.1: Surface numbering.

Note that in systems with reflectors, the thickness is usually negative to the next surface. This is because after a reflector, the next surface in the optical path is usually located in the negative Z direction from the reflecting surface. Thus, the thickness associated with a surface should not be thought of as an optical distance, but rather as what is the location on the Z axis of the next surface relative to that of the current surface.

The thickness associated with the image surface (THI SI) is unique. The actual image distance from the surface prior to the image surface (SI-1) to the image surface (SI) is the sum of the paraxial image distance and defocus term (THI SI). This is to accommodate the use of a paraxial image solve (PIM) plus a defocusing term. If the paraxial image solve is not used, the image surface thickness (THI SI) is automatically updated to show the difference to the paraxial focus.

There are two ways to enter and modify surface data. The first is the surface spreadsheet editor, which can be invoked from the *Edit* -> *Surfaces* menu or from the appropriate toolbar icon 🖆. The second is from the command line, which exists twice, under the main menu and as a floating dialog that can be placed anywhere on the screen.

#### 8.1 Surface Editor

The surface editor is a tabbed dialog which contains several spreadsheets for editing surface parameter from the graphical user interface (GUI). This allows entering surface (prescription) parameters solely

from the GUI, as an alternative to entering data on the command line (sect. 6). The surface editor is invoked from the main menu *Edit*  $\rightarrow$  *Surface Data* or by clicking on the icon in the toolbar or by entering EDI SUR in the command line. The surface parameter are grouped in several tabs as

📢 Su	rface Edi	tor: E:\optalix\ex	am	ples\Misc\DOU	BLE	_GAUSS-2.0TX							
Stand	lard Data	Decenter, Tilts A	sph	ere GRIN Sol	ves	Special Aperture	s	Hologram 🗍 I	Mis	c. Array			
	TYPE	Radius		Distance		GLASS		APE-Y	*.	Shape	Glb	THR	Comment 🔺
OBJ	S	0.0000000		0.1000000E+21				0.00	0	circular	0	0.00000	
1	S	31.9354000	۷	4.902000		LAK9		17.00	1	circular	0	0.00000	
2	S	95.0214000	۷	0.2260000				16.36	0	circular	0	0.00000	
3	S	18.9471000	۷	5.421000		LAK9		13.38	0	circular	0	0.00000	
4	S	51.7823000	۷	2.827000		SF8		12.29	0	circular	0	0.00000	
5	S	12.8019000	۷	6.849000				8.58	0	circular	0	0.00000	
STO	S	0.0000000		6.663000	۷			6.17	0	circular	0	0.00000	<b>_</b>
						·		-					▶
EFL =	FEL = 49.99958 BEL = 27.98572 FND = 2.500000 V PIM												
MAG	MAG = 0.000000 SYL = 37.53800 0AL = 65.45612 🔽 AF0												
Pos. 1 v Insert Surf. Insert File Delete Surf. Help Close													

Figure 8.2: Surface spreadsheet editor, invoked by the command EDI SUR.

## 8.2 Undo and Redo of Surface Parameter

It is possible to undo or redo virtually all parameter changes, including those entered from the various editors or from the command line. However, changes made to parameters from a macro, cannot be undone.

Undo is performed by clicking the left arrow symbol on the left side of the program main window, for a redo click on the corresponding right arrow symbol. The location of the toolbar containing the undo and redo symbols is shown in Fig. 8.3:



Figure 8.3: Undo and redo functions

From the command line, undo and redo is performed by the following commands:

UNDO	Undo a parameter change.
REDO	Redo a parameter change.

shown in Fig. 8.2):

# 8.3 Surface Parameters

The following table list the commands for defining or editing common lens parameter from the command line. The parameter of special surfaces, such as holograms, fresnel surfaces, decentered or tilted surfaces, are described in detail in the subsections to follow.

S rad thi gla	Shorthand entry, inserts a new surface at the current surface
	pointer. See also section 8.5 for a detailed explanation.
ASP [sij]	defines aspheric surface
SPH [sij]	defines spherical surface
NOR [sij]	defines "no-raytrace" surface
K [sij] value	conic constant
A [sij] value	$4^{th}$ order aspheric constant as defined in equation 8.1.
B [sij] value	$6^{th}$ order aspheric constant as defined in equation 8.1.
C [sij] value	$8^{th}$ order aspheric constant as defined in equation 8.1.
D [sij] value	$10^{th}$ order aspheric constant as defined in equation 8.1.
E [sij] value	$12^{th}$ order aspheric constant as defined in equation 8.1.
F [sij] value	$14^{th}$ order aspheric constant as defined in equation 8.1.
G [sij] value	$16^{th}$ order aspheric constant as defined in equation 8.1.
H [sij] value	$18^{th}$ order aspheric constant as defined in equation 8.1.
CON [sij]	defines conic surface
YTO	defines toric surface in Y
STO si	Makes surface i stop surface. The "s" qualifier is not manda-
STO i	tory. The following examples are equally valid: STO s3. STO
	3
	Surface type defined by a string, up to 6-characters long "cccccc". Examples:
SUT [sii] ABCD	SUT s1 AD: surface 1 is aspheric and decentered,
	SUT s23 si : surfaces 2 to 3 are spherical and gradient
	index.
	See also the list on available surface type qualifiers below (page
	68).
	Curvature pickup. Pick surfaces sij to surface sx. A neg-
	ative sign for sx picks the surface with opposite curvature.
CPI si.j sx	Example:
	cP1 S5 -5. curvature 5 is picked from surface 5 with oppo-
	Sitt Sigli.
	Distance pickup. Fick surfaces s1] to surface sx. A nega-
	Example:
DPI SI J SX	Example. DDL $c_{2}^{-3}$ : distance 5 is nicked from surface 3 with onno
	site sign
MDI ci i cy	Material nickup. The material properties of surface are are
INTI SI J SX	nicked up (copied) to surfaces si
TDI ci i cy	Tilt and decenter nickup. The tilt and/or decenter values are
	nicked up from surfaces si i Thus surfaces si i are
	tilted/decentered by the same amount than surface sy
	continued on next page

continued from previous page	
TPF si factor	Tilt/decenter pick-up factor. If factor is not 1.0, picked val- ues for tilts and decenters will be multiplied by factor
CUX [sij] curvature_x	Curvature in X/Z plane. This parameter is effective only for toric surfaces and requires the surface type "A" (aspheric).
CUY [sij] curvature_y	Curvature in Y/Z plane. This is the default for spherical sur- faces. See also the command RDY which specifies the radius instead of curvature.
CIY [sij] curvature_incr	Increment Y-curvature (CUY) immediately. Convenient for a power change to an unknown curvature value.
RDX [sij] radius_x	Radius in X/Z plane. This parameter is effective only for toric surfaces and requires the surface type "A" (aspheric).
RDY [sij] curvature_y	Radius in Y/Z plane. This is the default for spherical surfaces. See also the command CUY which specifies curvature instead of radius. Note: A radius value of 0 is not physically possible, and is therefore interpreted as a curvature of 0 (a flat surface).
THI [sij] [zij zk] thickness	Axial thickness (separation) from actual surface vertex to sub- sequent surface.
TIN [sij] thickness_incr	Increment distance (THI) immediately. Convenient for a change to an unknown thickness value.
THM [sij sk] mirr_thickness	Center thickness to back surface of first-surface mirror at surface sk respectively surfaces sij. Value is always positive.
THR [sij] reference_thickness	Axial separation of surface(s) ij to "referenced" surface. Used in conjunction with global referencing. This command must not be confused with THI (axial thickness). THR is re- ferred to a <i>preceding</i> surface whereas THI always refers to the <i>subsequent</i> surface. Thus, a referencing surface can have both THI and THR parameters. See also section 8.22 for a detailed explanation of the concept of global referencing. Note: Specify the referenced surface by the command GLB sij k
GRO [sij] ival	Grating order, an integer value. This command is obsolete, HOR should be used instead.
HOR [sij] ival	Hologram diffraction order, an integer value.
GRX [sij] grating_freq_x	Grating frequency in grooves/mm (grooves parallel to X-axis)
GRY [sij] grating_freq_y	Grating frequency in grooves/mm (grooves parallel to Y-axis)
NSS [sij]	Make the surface(s) sij non-sequential.
MXH [sij] n_hits	Maximum number of allowable ray hits at non-sequential sur- face (default : n_hits = 10)
	continued on next page

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REFL [sij]	Reflect all rays (mirror surface).
REFR [sij]	Refract all rays. Total internal reflection (TIR) is a failure.
TIR [sij]	Total internal reflection. This surface acts like a mirror surface (REFL) except that rays that do not satisfy TIR condition are reported as failure.
RMD [sij] REFR REFL TIR	Refractive/reflective mode. Available modes are REFR = refract all rays at surface(s) sij = default mode. REFL = reflect all rays at surface(s) sij TIR = only reflects rays obeying TIR condition This command complements the explicit commands REFR, REFL and TIR as given above.
MFL si module_efl	Module focal length. si is the first surface of the module range.
SPG [sij sk] spec_gravity	Specific gravity in $g/cm^3$ . Value is taken from glass catalogue but may be overwritten by the SPG command.

## 8.4 Infinity Values

Because infinity values cannot be accurately represented in computers, the following conventions apply:

**Distances, Separations:** Any distance greater than  $10^{10}$  is considered as an infinite value. This convention particularly applies to object distances at infinity. Make sure that the object distance (THI  $\pm 0$ ) is  $> 10^{10}$  to ensure infinitely distant objects.

**Radius, Curvature:** Any radius greater  $10^{10}$  is considered as infinity, that is, the surface is assumed perfectly flat. A special case is the surface radius 0, for example RDY sk 0. This command automatically defaults to a flat surface with infinite surface radius (curvature = 0, i.e. CUY sk 0).

# 8.5 Surface Shorthand Entry

A shorthand entry of a spherical surface is obtained by the command:

```
S rad_curv thickness glassname
```

where

rad_curv	is the radius or curvature in Y-direction. Radius or curvature entry is defined
	by the RDM command (see section 7.1 page 43),
thickness	is the axial separation right of the surface vertex
glassname	is the glass manufacturer's designation

The default surface type on surface shorthand entry is spherical.

# 8.6 Surface Type

Surface types are characterized by six-character strings which are assigned to each surface. The surface type is defined by the following command:

SUT si..j cccccc

where cccccc is an arbitrary sequence of surface descriptors ( a character). Surface types are categorized into obligatory and optional ones, according to the following table.

	<b>Obligatory Surface Types</b>	0	ptional Surface Types, in arbitrary order
S	Spherical surface	D	Decentered and/or tilted surfaces
A	Aspheric surface, see sections 8.7.1 to 8.7.5.	M	Mirror
L	Lens module (ideal lens)	G	Grating surface
X	"No-raytrace" surface. Only transforms sur- face coordinates without actually tracing rays to this surface. See sect. 8.23	Н	Holographic surface
U	User-defined surface	F	Fresnel Surface
		Ι	Gradient index (GRIN) surface
		N	Non-sequential surface (NSS), must be used in combination with surface type "D"
		Р	Pipe, (Light Pipe, step index fiber). The cone angle of tapered pipes/fibers is defined by the semi-apertures of the end surfaces
		R	Array (Lens Array)
		Т	Total internal reflection (TIR) surface (see sect. 8.13, page 98)
		Z	Zernike surface
		C	Radial Spline deformation
		W	2-dimensional surface deformation, given as gridded data
		E	pure 2-dimensional spline (non- symmetric), no base surface. In preparation.

One of the obligatory surface types ("A", "S", "X", "U" or "L") must always be specified. "A" and "S" describe the base surface (aspheric or spherical). Surface type "L" (lens module) does not specify a base surface, since it only has transformational properties. "L" is also an exception of the rule, because no optional surface types are allowed in addition to the "L" character.

Optional surface descriptors may be arbitrarily combined in order to build complex surfaces. For example,

SUT s1..3 DAM sets the surface type of the surfaces 1 - 3 to D = decentered, A = aspheric, M = mirror

The order of surface type qualifiers does not matter, i.e.

SUT s1..3 DAM SUT s1..3 AMD SUT s1..3 MDA

are equivalent.

**Note:** Gradient index surfaces and step index fibers require two qualifiers, one to define the surface type and a second one for the material properties (GRIN or step index). For example,

- SI denotes a spherical surface with gradient index material attached,
- SP is a spherical surface with step index properties.

## 8.7 Aspheric Surfaces

Aspheric surfaces are commonly defined by polynomial expressions in one dimension which are then rotated about the local Z-axis to form the surface. The following types of polynomial aspheres are available:

- even power polynomial asphere, up to  $18^{th}$  order,
- odd power polynomial asphere, up to  $9^{th}$  order,
- odd power special polynomial asphere, up to  $30^{th}$  order,
- XY polynomial surface, up to  $10^{th}$  order.
- anamorphic (biconic) surface, up to  $10^{th}$  order,
- toroidal surface,
- cylindrical surface.
- Qcon polynomial
- Qbf polynomial
- Xfreeform asphere, a combination of anamorphic, even and XY polynomial asphere, plus standard Zernike coefficients.

Aspheric surfaces are defined by a type designator command ASP sk or by changing the surface type to "A". The surface form is further defined by coefficients of various types.

Aspheric surfaces command overview:

A	SP sij sk EVEN ODD9 ODD30 XYP  AAS CYL QCN QBF XFF								
	Converts surface(s) sij sk to type aspheric. Any corresponding coeffi-								
	cients are appropriately converted. A warning message is issued if the order								
	of coefficients does not match. For example, an ASP EVEN type asphere								
	can be converted to an ASP ODD30 asphere, whereas the inverse conver-								
	sion (ASP ODD30 to ASP EVEN) may result in loss of coefficients because								
	odd power coefficients cannot be modelled in the ASP EVEN type surface.								
	See also the ATY command below.								
A	TY sij sk EVEN ODD9 ODD30 XYP  AAS CYL QCN QBF XFF								
	Only changes asphere type without converting coefficients. The type of of								
	higher order polynomials is defined as:								
	EVEN = only even power polynomial according to Eq. $8.1$ ,								
	ODD9 = mixed odd and even powers according to Eq. $8.5$ .								
	ODD30 = extended odd and even powers,								
	XYP = XY polynomial up to $10^{th}$ order,								
	AAS = anamorphic asphere (biconic in absence of higher-order coefficients).								
	QBF = Qbfs aspheric surface.								
	QCN = Qcon a spheric surface.								
	CYL = cylindrical surface.								
	XFF = Xfreeform surface								
	Note that the coefficients for the even and odd9 asphere types are entered								
	by the A, B, C, D, E, F, G, H commands, whereas the coefficients for the								
	ODD30 and XYP asphere types must be entered using the SCO command								
	(see below). Alternatively, a dialog-based entry is provided by the EDI SPS								
	command.								

Code V compatibility commands				
	Change surface profile to ODD, XYP, QCN or QBF special as-			
	pheric surface. Automatically sets surface type to "A" and asphere			
	type according to the equivalences			
	ATY odd30 for SPS ODD			
	ATY xyp for SPS XYP.			
	SPS surface profile is determined by the curvature (RDY or CUY)			
SPS ODD XYP QCN QBF	and the SCO coefficients. If the surface is changed from an as-			
XFF   ZFR   ZFE   ZRN	pheric surface of kind "EVEN" or "ODD9" to an SPS surface,			
sij sk	then any corresponding surface parameters are retained and stored			
	in the appropriate SCO coefficients. All other SCO coefficients			
	are set to zero.			
	ZFR   ZFE   ZRN : Enables Zernike coefficients at surface range			
	sij sk. For details see ZTYP command, (page 149).			
SCO sij sk ci				
coefficient	Coefficients for describing the SPS ODD XYP QCN QBF			
	surface(s) sij sk. The coefficients differ in meaning for			
	each ODD   XYP type as described in sections 8.7.4 and 8.7.5			
	respectively.			
continued on next page				

continued from previous page		
YTO sij sk	Defines a Y-toroid. The surface can be an ODD9 or EVEN power asphere in the Y-plane but is always assumed spherical in the X-plane. The Y-toroid degenerates to a sphere for $CUX =$ CUY (respectively $CUX = 0$ ) and $K = A = B = C = D = E = F =G = H = 0$ .	
CYL sij sk	Defines a cylinder. For details see sect. 8.7.7 (page 78).	
IC sk sii Yes No	Intersection direction. As there may be more than one intersection of a ray with a surface, this option allows choosing the alternate intersection point from the one normally used. This option is nor- mally not needed except when rays are at high angle to the local surface axis.	
	<pre>IC Yes = default, IC No = selects alternate intersection point.</pre>	
	In the surface editor, IC can be set in the "Misc" tab.	
	See also the notes on alternate intersection points in sect. 8.8.	

Note that aspheric surfaces always require the surface type (SUT) "A", which must replace the surface types "S", "L", "U" or "X". For example, simultaneous specification of surface types "SA", "LA" or "XA" is not permitted. See also a detailed description of surface types in section 8.6 on page 68.

#### 8.7.1 "EVEN" Power Asphere

The "EVEN" power polynomial aspheric surface is defined as

$$z = \frac{ch^2}{1 + \sqrt{1 - (K+1)c^2h^2}} + A \cdot h^4 + B \cdot h^6 + C \cdot h^8 + D \cdot h^{10} + E \cdot h^{12} + F \cdot h^{14} + G \cdot h^{16} + H \cdot h^{18}$$
(8.1)

where:  $\begin{cases} c = \text{vertex curvature (in } mm^{-1}) \\ K = \text{conic constant} \\ A, B, C, D, E, F, G, H = \text{asph. coefficients} \\ h^2 = x^2 + y^2 (\text{in mm}) \\ x, y = \text{surface coordinates (in mm)} \end{cases}$ 

The EVEN power asphere is a rotationally symmetric surface, that is, the conic/polynomial profile defined in Eq. 8.1 is rotated about the local Z-axis.

The conic constant K describes surfaces of conic sections:

		K	<	-1	Hyperbola
		K	=	-1	Parabola
-1	<	K	<	0	Ellipse at major axis (prolate ellipse)
		K	>	0	Ellipse at minor axis (oblate ellipse)
		K	=	0	Sphere

Table 8.4: Geometric interpretation of conic constant K
A different variant of equation 8.1 is occasionally in use:

$$z = \rho h^2 / \left( 1 + \sqrt{1 + (1 - \kappa \rho^2 h^2)} \right) + A \cdots h^4 + B \cdots h^6 + \cdots$$
 (8.2)

Since both, K and  $\kappa$ , are termed conic constants and both equations are of similar form, they can be easily confused. For the sake of clarity, equation 8.1 is used consistently in OpTaliX. The numerical eccentricity  $\varepsilon$  and the conic constant k are then related by:

$$K = -\varepsilon^2 \quad \text{ellipse at major axis} \tag{8.3}$$

$$\frac{K}{K+1} = \varepsilon^2 \quad \text{ellipse at minor axis} \tag{8.4}$$

Equation 8.3 is also valid for a hyperbola.



Figure 8.4: Conic sections of aspheric surfaces.

#### 8.7.2 "ODD9" Power Asphere

The difference between this surface and the "EVEN" power polynomial asphere defined in the previous section is the form of the expansion polynomial, which includes both the odd and even powers of radial distance up to  $9^{th}$  order. In addition, the terms start at power 2 instead at power 4.

$$z = \frac{ch^2}{1 + \sqrt{1 - (K+1)c^2h^2}} + A \cdot h^2 + B \cdot h^3 + C \cdot h^4 + D \cdot h^5 + E \cdot h^6 + F \cdot h^7 + G \cdot h^8 + H \cdot h^9$$
(8.5)

The  $A \cdot h^2$  term is taken into account in paraxial calculations. The quadratic term describes a parabola with vertex curvature  $2 \cdot A$ . Thus, the effective curvature used in paraxial analysis is  $c = c_o + 2 \cdot A$ . The ODD power asphere is a rotationally symmetric surface, that is, the conic/polynomial profile defined in Eq. 8.5 is rotated about the local Z-axis.

## 8.7.3 Ellipse at major or minor Axis in the EVEN and ODD9 Asphere Models

The terminology "ellipse at major respectively minor axis" as used in the previous sections often leads to confusion. The EVEN and ODD9 asphere surfaces are primarily rotationally symmetric surfaces, if we assume  $c_x = CUX = 0$  (special case of toric surface). That is, the surface is generated by rotating a 2-dimensional curve (conic or polynomial) in the Y/Z-plane about the local Z-axis.

This concept is important to understanding how elliptical surfaces are formed in the EVEN and ODD9 asphere models. Eqs. 8.1 and 8.5 only define the sag in the Y/Z-plane. Rotating these curves about the local Z-axis describes an ellipsoid for -1 < K < 0 (ellipse at major axis), however, it does NOT for elliptical sections at the minor axis (K > 0).

Figures 8.5 and 8.6 illustrate the difference.



Figure 8.5: Definition of an elliptical section at the major axis (-1 < K < 0). Left: Section of the ellipse. Right: Perspective view showing the resulting surface.



Figure 8.6: Definition of an elliptical section at the minor axis (K > 0). Left: Section of the ellipse. Right: Perspective view showing the resulting surface.

Thus, an elliptical section defined at the minor axis does not describe a "true" ellipsoid with its minor axis aligned with the local Z-axis. If you need to model a true ellipsoid aligned at the minor axis, use the anamorphic (biconic) surface model as described in section 8.7.6.

## 8.7.4 "ODD30" Power Asphere

The "ODD30" asphere is an extension of the "ODD9" surface to  $30^{th}$  order including both odd and even powers of radial distance. It is a purely rotationally symmetric surface. Due to the larger number

of coefficients accepted, it is handled as a *special* aspheric surface respectively SPS in the Code V lingo. Basically, a *special* surface (SPS) is handled like a "user defined surface" (UDS) because it uses the same domain of coefficients. The only difference between the two variants is that special surface coefficients are entered by the SCO command and user defined surface coefficients are entered by the UCO command. User defined surfaces and special surfaces are distinguished by the surface type

- for special surfaces (of kind EVEN, ODD9, ODD30, XYP) А
- for user defined surfaces U

$$z = \frac{ch^2}{1 + \sqrt{1 - (K+1)c^2h^2}} + C_2 \cdot h + C_3 \cdot h^2 + C_4 \cdot h^3 + C_5 \cdot h^4 + C_6 \cdot h^5 + \cdots + C_{31} \cdot h^{30}$$
(8.6)

where:  $\begin{cases} c = \text{vertex curvature (in } mm^{-1}) \\ K = \text{conic constant} \\ C_i = \text{coefficient of } h^{i-1}, \text{ for } 2 \le i \le 31 \\ h^2 = x^2 + y^2 \text{ (in mm)} \\ x, y = \text{surface coordinates (in mm)} \end{cases}$ 

If all  $C_i$  coefficients are zero (the default), a pure conic surface results. The maximum number of terms to use in the expansion can be specified with coefficient  $C_{32}$  (C32) in order to speed up computation. If C32 is 0, then all 31 coefficients are used.

The table below gives the coefficient numbers for the surface parameters of the ATY ODD30 asphere type (use alternatively SPS ODD command).

Coefficient	Definition
C1	Conic constant
C2	1 <sup>st</sup> order aspheric coefficient
C3	$2^{nd}$ order aspheric coefficient
C4	$3^{rd}$ order aspheric coefficient
C5	4 <sup>th</sup> order aspheric coefficient
C6	$5^{th}$ order aspheric coefficient
C7	6 <sup>th</sup> order aspheric coefficient
C8	7 <sup>th</sup> order aspheric coefficient
C9	$8^{th}$ order aspheric coefficient
C10	9 <sup>th</sup> order aspheric coefficient
C11	10 <sup>th</sup> order aspheric coefficient
C12	11 <sup>th</sup> order aspheric coefficient
C13	12 <sup>th</sup> order aspheric coefficient
C14	13 <sup>th</sup> order aspheric coefficient
C15	14 <sup>th</sup> order aspheric coefficient
÷	÷
C31	$30^{th}$ order aspheric coefficient
C32	Number of terms to use in the expansion

Entering coefficients C1 to C32 is accomplished by the SCO command explained on page 82.

In the surface editor the SPS ODD surface is selected from the 'Asph.Type' column in the 'Asphere' tab. Use the pull-down menu to define the proper asphere type, as shown in Fig. 8.7.

Note that the K, A, B, C, ... columns are greyed out as they have no meaning for SPS ODD surfaces. Instead, invoke the SPS/UDS editor to edit ODD/ODD30 coefficients. This is performed from the main menu *Edit -> SPS/UDS Coefficients* or from the command line by entering EDI UDS

📢 Surface Editor: E:\optalix\examples\Misc\DOUBLE_GAUS5.0TX								×			
Standard Dat	a Decenter, Ti	ilts A	Asphere GRIN :	So	lves   Special Ape	rtur	res Hologram M	isc			
	Asph.Type	Pik	K (Conic Const.)		A		B		С		
OBJ S	even, 18th ord		0.000000		0.000000		0.0000000		0.0000000	Τ	
1 A	odd 30th o 💌		0.000000		0.0000000		0.0000000		0.0000000		
2 S	even, 18th ord		0.000000		0.0000000		0.0000000		0.0000000	Τ	
3 S	odd, 9th order odd 30th order		0.000000		0.0000000		0.0000000		0.0000000	Τ	-
4	XY polynomial									Þ	

Figure 8.7: Defining SPS ODD aspheric surfaces.

### 8.7.5 "XY" Polynomial Asphere

The XY polynomial asphere is a  $10^{th}$  order polynomial surface added to a base conic. The polynomial is expanded into monomials of  $x^m y^n$ , where  $m + n \le 10$ . The equation is

$$z = \frac{ch^2}{1 + \sqrt{1 - (K+1)c^2h^2}} + \sum_{i=2}^{66} C_i x^m y^n$$
(8.7)

where:  $\begin{cases} c = \text{vertex curvature (in } mm^{-1}) \\ K = \text{conic constant} \\ C_i = \text{coefficient of the monomial } x^m y^n \\ h^2 = x^2 + y^2 \text{ (in mm)} \\ x, y = \text{surface coordinates (in mm)} \end{cases}$ 

The maximum number of terms used in the expansion can be specified with C67, which speeds up computation. If C67 is 0, all 66 terms are used.

Coefficient	Definition	Coefficient	Definition
C1	Conic constant	C34	$x^2y^5$
C2	x	C35	$xy^6$
C3	y	C36	$y^7$
C4	$x^2$	C37	$x^8$
C5	xy	C38	$x^7y$
C6	$y^2$	C39	$x^{6}y^{2}$
C7	$x^3$	C40	$x^5y^3$
C8	$x^2y$	C41	$x^4y^4$
C9	$xy^2$	C42	$x^{3}y^{5}$
C10	$y^3$	C43	$x^2y^6$
C11	$x^4$	C44	$xy^7$
C12	$x^3y$	C45	$y^8$
C13	$x^2y^2$	C46	$x^9$
C14	$xy^3$	C47	$x^8y$
C15	$y^4$	C48	$x^7y^2$
C16	$x^5$	C49	$x^{6}y^{3}$
C17	$x^4y$	C50	$x^{5}y^{4}$
C18	$x^3y^2$	C51	$x^{4}y^{5}$
C19	$x^2y^3$	C52	$x^{3}y^{6}$
C20	$xy^4$	C53	$x^2y^7$
		С	ontinued on next page

C21	$y^5$	C54	$xy^8$
C22	$x^6$	C55	$y^9$
C23	$x^5y$	C56	$x^{10}$
C24	$x^4y^2$	C57	$x^9y$
C25	$x^3y^3$	C58	$x^8y^2$
C26	$x^2y^4$	C59	$x^7y^3$
C27	$xy^5$	C60	$x^6y^4$
C28	$y^6$	C61	$x^5y^5$
C29	$x^7$	C62	$x^4y^6$
C30	$x^6y$	C63	$x^3y^7$
C31	$x^5y^2$	C64	$x^2y^8$
C32	$x^4y^3$	C65	$xy^9$
C33	$x^3y^4$	C66	$y^{10}$
		C67	Number of terms

Entering coefficients C1 to C67 is accomplished by the SCO command explained on page 82. In the surface editor the SPS XYP surface is selected from the 'Asph.Type' column in the 'Asphere'

tab. Use the pull-down menu to define the proper asphere type, as shown in Fig. 8.8.

Sunace	concorre: (opcal	in (e	kamples (Misc (D		DDLC_GAUSS.017	~				•
Standard Da	ta Decenter, Ti	ilts /	Asphere GRIN	So	lves   Special Aper	tur	es Hologram Mi	sc.		
	Asph.Type	Pik	K (Conic Const.)		. Α		В		С	
DBJ S	even, 18th ord		0.0000000	Γ	0.0000000		0.0000000	Т	0.000000	T
1 A	XY polynor 💌		0.000000		0.0000000		0.0000000		0.000000	
2 S	even, 18th ord		0.000000	Γ	0.0000000		0.0000000	Τ	0.000000	
3 S	odd, 9th order		0.000000		0.0000000		0.0000000		0.0000000	

Figure 8.8: Defining SPS ODD or SPS XYP aspheric surfaces. Note that the K, A, B, C, ... coefficients are greyed out and cannot be edited in the surface editor. For editing SPS ODD or SPS XYP coefficients, use the EDI UDS command.

Note that the K, A, B, C, ... columns are greyed out as they have no meaning for SPS ODD or SPS XYP surfaces. Instead, invoke the SPS/UDS editor to edit XYP coefficients. This is performed from the main menu *Edit -> SPS/UDS Coefficients* or from the command line by entering EDI UDS

### 8.7.6 Anamorphic (Biconic) Asphere

The anamorphic asphere surface exhibits bilateral symmetry in both sections X and Y. The equation is:

$$z = \frac{c_x x^2 + c_y y^2}{1 + \sqrt{1 - (1 + K_x) c_x^2 x^2 - (1 + K_y) c_y^2 y^2}} + A_R \left[ (1 - A_P) x^2 + (1 + A_P) y^2 \right]^2 + B_R \left[ (1 - B_P) x^2 + (1 + B_P) y^2 \right]^3 + C_R \left[ (1 - C_P) x^2 + (1 + C_P) y^2 \right]^4 + D_R \left[ (1 - D_P) x^2 + (1 + D_P) y^2 \right]^5$$

$$(8.8)$$

Variable	Command	Description
Z	SAG	the sag of the surface at the local surface coordinates
$c_x, c_y$	CUX, CUY	the curvatures in X and Y
$K_x, K_y$	КХ, КҮ	conic constants in X and Y. The definition of $K_y$ is equivalent to the conic constant K as given in table 8.4 (page 71).
$A_R$	AR	rotationally symmetric coefficient, 4 <sup>th</sup> order
$B_R$	BR	rotationally symmetric coefficient, 6 <sup>th</sup> order
$C_R$	CR	rotationally symmetric coefficient, $8^{th}order$
$D_R$	DR	rotationally symmetric coefficient, $10^{th} order$
$A_P$	AP	non-rotationally symmetric coefficient, $4^{th}order$
$B_P$	BP	non-rotationally symmetric coefficient, 6 <sup>th</sup> order
$C_P$	CP	non-rotationally symmetric coefficient, 8 <sup>th</sup> order
$D_P$	DP	non-rotationally symmetric coefficient, $10^{th} order$

where:

Note that the anamorphic surface reduces to the standard EVEN power asphere (see sect. 8.7.1) when

Variables	Commands
$c_x = c_y$	CUX = CUY
$k_x = k_y$	КХ <b>=</b> КҮ
$A_P = B_P = C_P = D_P = 0$	AP = BP = CP = DP = 0

	Specifies anamorphic asphere. Parameters are
	X-Curvature/X-Radius (CUX/RDX),
	Y-Curvature/Y-Radius (CUY/RDY),
	X-conic constant (KX),
AAS sk sij	Y-conic constant (KY),
	$4^{th}-10^{th}$ order rotationally symmetric coefficients (AR,
	BR, CR, DR),
	$4^{th} - 10^{th}$ order non-rotationally symmetric coefficients
	(AP, BP, CP, DP).
ATY sk sij AAP	as above, sets asphere type (ATY) to anamorphic asphere
KX sk sij	X-conic coefficient
X_conic_const	
KY sk sij	Y-conic coefficient, identical with K
Y_conic_const	
AR sk sij coeff	4 <sup>th</sup> order rotational symmetric coefficient
BR sk sij coeff	6 <sup>th</sup> order rotational symmetric coefficient
CR sk sij coeff	8 <sup>th</sup> order rotational symmetric coefficient
DR sk sij coeff	$10^{th}$ order rotational symmetric coefficient
AP sk sij coeff	4 <sup>th</sup> order non-rotational symmetric coefficient
BP sk sij coeff	6 <sup>th</sup> order non-rotational symmetric coefficient
CP sk sij coeff	8 <sup>th</sup> order non-rotational symmetric coefficient
DP sk sij coeff	10 <sup>th</sup> order non-rotational symmetric coefficient

# **Commands:**

# 8.7.7 Cylindrical Surfaces

A cylinder surface is defined by CUX/RDX or CUY/RDY, depending on the orientation of the cylinder. By default, the axis of the cylinder is assumed along the X-axis (that is, CUY/RDY  $\neq 0$ , CUX/RDX = 0). For arbitrary orientations of the cylinder axis use  $\gamma$ -rotation (CDE).

CYL sk sij	Defines cylinder surface. By default, the cylinder axis is assumed
	along the local X-axis, i.e. $CUY/RDY \neq 0$ , $CUX/RDX = 0$ . The
	profile in the local Y/Z-section can be a sphere or an EVEN as-
	phere whereas in the local X/Z-plane only spherical sections are
	allowed (See also toroidal surfaces, page 78 with the cylinder sur-
	face as special case). Use $\gamma$ -rotation (CDE) for arbitrary orienta-
	tion of the cylinder axis.
ASP CYL sk sij	As above. Complementary syntax.

## Notes:

- Cylinder surfaces may also be defined using the regular EVEN or ODD9 asphere types. In this case, CUX/RDY ≠ 0 defines a toroidal surface, which, for very large radii (RDX > 10<sup>10</sup>), very well approximates a plane section in X.
- In the Y/Z-section any profile according to the EVEN asphere type (see Eq. 8.1, page 71) is allowed, whereas in the X/Z-section the profile is a straight line. Use  $\gamma$ -rotation (CDE) for any other orientation of the cylinder axis.

# Examples:

Cylinder axis along X-axis:	CYL sl	
	RDY s1 1	00
	<b>1</b>	
Cylinder axis along Y-axis:	CYL sl	
	RDX s1 1	00
Arbitrary cylinder orientation :	CYL sl	
	RDY s1 1	00
	CDE s1 4	5 ! $\gamma$ -rotation 45°

Notice that cylinder surfaces may also be defined using the regular EVEN or ODD9 asphere types (see sect. 8.7.1 and 8.7.2). In this case, CUX/RDX  $\neq 0$  defines a toroidal surface, which, for very large radii (RDX  $\geq 10^{10}$ ), very well approximates a plane section in X.

# 8.7.8 Toroidal Surfaces

Toroidal surfaces exhibit different radii/curvatures in X- and Y-direction. A toroidal surface is a subset of the general aspheric surface (type EVEN or ODD9, see sections 8.7.1 and 8.7.2) and is distinguished from a rotationally symmetric asphere by a non-zero X-curvature ( $CUX \neq 0$ ). Toroidal surfaces must be of surface type "A" (asphere). Commands for entering curvatures in X-plane and Y-plane are:

! curvature in X-direction	curv	sij	CUX
! radius in X-direction	radius	sij	RDX
! curvature in Y-direction	curv	sij	CUY
! radius in Y-direction	radius	sij	RDY

Toroidal surfaces are described by the following extension to the aspheric equation 8.1:

$$z = F(y) + \frac{c_x}{2} \left( x^2 + z^2 - F(y)^2 \right)$$
(8.9)

where  $c_x$  is the curvature in the X/Z plane and F(y) is equivalent to equation 8.1 respectively 8.5. Equation 8.9 can be transformed to the normal form by:

$$0 = x^{2} - \left(F(y)^{2} - \frac{2}{c_{x}}F(y)\right) + z^{2} - \frac{2}{c_{x}}z + \frac{1}{c_{x}^{2}} - \frac{1}{c_{x}^{2}}$$
(8.10)

$$0 = x^{2} - \left(F(y) - \frac{1}{c_{x}}\right)^{2} + \left(z - \frac{1}{c_{x}}\right)^{2}$$
(8.11)

thus, the toric deformation of the aspheric surface in the X/Z plane can be a sphere only. The aspheric deformations in the Y/Z plane remain as described in equations 8.1 and 8.5.

The cylinder surface is a special case of the toroidal surface with  $\rho_x = 10^{-10}$ . While the EVEN/ODD surface is more general, there is a special asphere type "CYLINDER" (page 78) which simplifies data input for this special surface/asphere type.

#### 8.7.9 Q-Type Polynomials

Aspheric surfaces using Q-type polynomials as described by G.Forbes [63, 64] offer several advantages over the classical monomials as given in sect. 8.7.1. Major advantages are:

- The coefficients have a physical meaning. In particular, Q-type polynomials for aspheric surfaces have units of length and their value directly expresses their contribution to the surface departure.
- The polynomial terms form a descending series giving a clear indication as to when a coefficient becomes irrelevant.
- Q-type polynomial coefficients can be given meaningful tolerances for the fabricator.
- The aspheric terms are orthogonal (within a normalization radius). Each term is unique and simplifies tolerancing.
- Easier definition of slope constraints for improvement of manufacturability.
- Fewer digits of precision are required. This simplifies the numerical burden for transferring asphere prescription data to optical fabrication.
- Helps to reduce the number of terms.

Two Q-type polynomial descriptions are available:

- The Qbfs ("best fit") polynomial form is characterized by an RMS slope departure from a bestfit sphere. The RMS slope of the departure provides a sensible metric of the testability of the surface. It can easily be calculated from the Qbfs coefficients, and it is proportional to mean fringe density. Typically it is intended for use with "mild" aspheres.
- The Qcon ("conic") form is characterized by the sag departure from a base conic.

# 8.7.10 Qbfs Polynomial (SPS QBF)

The SPS QBF surface describes symmetrical aspheres using Qbfs polynomials up to  $30^{th}$  order. The aspheric deviation is defined an the basis of a best-fit sphere. The surface sagitta is defined by

$$z = \frac{c_{bfs}r^2}{1 + \sqrt{1 - c_{bfs}^2 \cdot r^2}} + \frac{u^2(1 - u^2)}{\sqrt{1 - c_{bfs}^2 r_n^2 u^2}} \sum_{m=0}^{13} a_m Q_m^{bfs}(u^2)$$
(8.12)

with

z sag of the surface perpendicular to the vertex tangent plane (parallel to the local z-axis)

 $c_{bfs}$  curvature of best-fit sphere

 $r = \sqrt{x^2 + y^2}$  radial distance from vertex

$$r_n$$
 normalization radius.  
 $u = r/r_n$ 

 $a_m = m^{th}Q^{bfs}$  coefficient

 $Q_m^{bfs}$  the  $Q^{bfs}$  polynomial of order m.

Given the relation  $u^4 \cdot u^{2m} = u^{2m+4}$ , the order of the  $Q^{bfs}$  polynomial is 2m + 4. The range 0-13 for m yields orders 4-30.

In explicit notation, the first six Qbfs basis elements are:

Term	Qbfs polynomial expression
1	1
2	$\left  \frac{1}{\sqrt{19}} \left( 13 - 16u^2 \right) \right $
3	$\sqrt{\frac{2}{95}} \left[ 29 - 4x \left( 25 - 19u^2 \right) \right]$
4	$\left[\sqrt{\frac{2}{2545}} \left\{207 - 4u^2 \left[315 - u^2 \left(577 - 320u^2\right)\right]\right\}\right]$
5	$\left  \frac{1}{3\sqrt{131831}} \left( 7737 - 16u^2 \left\{ 4653 - 2u^2 \left[ 7381 - 8u^2 \left( 1168 - 509u^2 \right) \right] \right\} \right) \right.$
6	$\left  \frac{1}{3\sqrt{6632213}} \left[ 66657 - 32u^2 \left( 28338 - u^2 \left\{ 135325 - 8u^2 \left[ 35884 - u^2 \left( 34661 - 12432u^2 \right) \right] \right\} \right) \right]$

The table below lists the coefficient numbers for the surface parameters of the SPS QBF asphere type. (use alternatively ATY QBF command).

Coefficient	Definition	
C1	Conic constant	
C2	Normalization radius (NRAD). If a normalization radius is not defined, the	
	clear Y semi-aperture (e.g. CIR, REY, etc.) is used instead.	
C3	$4^{th}$ order Qbfs coefficient ( $a_0$ )	
C4	$6^{th}$ order Qbfs coefficient ( $a_1$ )	
C5	$8^{th}$ order Qbfs coefficient ( $a_2$ )	
C6	$10^{th}$ order Qbfs coefficient ( $a_3$ )	
C7	$12^{th}$ order Qbfs coefficient ( $a_4$ )	
C8	$14^{th}$ order Qbfs coefficient ( $a_5$ )	
C9	$16^{th}$ order Qbfs coefficient ( $a_6$ )	
C10	$18^{th}$ order Qbfs coefficient ( $a_7$ )	
C11	$20^{th}$ order Qbfs coefficient ( $a_8$ )	

continued on next page

C12	$22^{th}$ order Qbfs coefficient ( $a_9$ )
C13	$24^{th}$ order Qbfs coefficient ( $a_{10}$ )
C14	$26^{th}$ order Qbfs coefficient ( $a_{11}$ )
C15	$28^{th}$ order Qbfs coefficient ( $a_{12}$ )
C16	$30^{th}$ order Qbfs coefficient ( $a_{13}$ )
	••••
C32	Number of terms to use in the expansion ( $\frac{1}{6}2$ , $\frac{1}{13}$ ). If zero (0),
	OpTaliX automatically determines the number of terms by searching for the
	highest order non-zero coefficient.

Entering coefficients C1 to C32 is accomplished by the SCO command, explained in general on page 82. Specifically for Qbfs surfaces the necessary commands are:

SPS QBF sij sk	Change surface profile to QBF special aspheric surface.
	Defines coefficients for SPS QBF surface(s) sij sk. If more
SCO si isk ci i	than one coefficient is entered, all coefficients must be specified
coefficient(s)	on the same command line. Example:
	SCO s3 c35 0.1 0.2 0.3

# 8.7.11 Qcon Polynomial (SPS QCN)

The SPS QCN surface describes symmetrical aspheres using Qcon polynomials as described by Forbes [63] up to  $30^{th}$  order. The aspheric deviation is defined an the basis of a base conic. The surface sagitta is defined by

$$z = \frac{c \cdot r^2}{1 + \sqrt{1 - (1 + k)c^2r^2}} + u^4 \sum_{m=0}^{13} a_m Q_m^{con}(u^2)$$
(8.13)

with

zsag of the surface perpendicular to the vertex tangent plane (parallel to the local z-axis)cvertex curvature (CUY)kconic constantr $= \sqrt{x^2 + y^2}$  radial distance from vertex $r_n$ normalization radius (NRAD).

$$u = r/r_n$$

$$a_m \qquad m^{th}Q^{con}$$
 coefficient

 $Q_m^{con}$  the  $Q^{con}$  polynomial of order m.

The Q vector at a particular  $x = u^2$  is calculated by the following recurrance relationship:

$$Q(0,x) = 1$$

$$Q(1,x) = 6x - 5$$

$$Q(n,x) = \frac{(2*n+3)((n+1)(n+2)(2x-1) - 4)Q(n-1,x) - (n-1)(n+2)(n+3)Q(n-2,x))}{n(n+1)(n+4)}$$

In explicit notation, the first six Qcon basis elements are:

81

1	1
2	$6u^2 - 5$
3	$15 - 14u^2(3 - 3u^2)$
4	$-\left\{35 - 12u^{2}\left[14 - u^{2}\left(21 - 10u^{2}\right)\right]\right\}$
5	$70 - 3u^2 \left\{ 168 - 5u^2 \left[ 84 - 11u^2 \left( 8 - 3u^2 \right) \right] \right\}$
6	$-\left[126 - u^{2} \left(1260 - 11u^{2} \left\{420 - u^{2} \left[720 - 13u^{2} \left(45 - 14u^{2}\right)\right]\right\}\right)\right]$

The table below lists the coefficient numbers for the surface parameters of the SPS QCN asphere type. (use alternatively ATY QCN command).

Definition	
Conic constant	
Normalization radius (NRAD). If a normalization radius is not defined, the	
clear Y semi-aperture (e.g. CIR, REY, etc.) is used instead.	
$4^{th}$ order Qcon coefficient $(a_0)$	
$6^{th}$ order Qcon coefficient $(a_1)$	
$8^{th}$ order Qcon coefficient $(a_2)$	
$10^{th}$ order Qcon coefficient ( $a_3$ )	
$12^{th}$ order Qcon coefficient ( $a_4$ )	
$14^{th}$ order Qcon coefficient ( $a_5$ )	
$16^{th}$ order Qcon coefficient ( $a_6$ )	
$18^{th}$ order Qcon coefficient ( $a_7$ )	
$20^{th}$ order Qcon coefficient ( $a_8$ )	
$22^{th}$ order Qcon coefficient ( $a_9$ )	
$24^{th}$ order Qcon coefficient ( $a_{10}$ )	
$26^{th}$ order Qcon coefficient ( $a_{11}$ )	
$28^{th}$ order Qcon coefficient ( $a_{12}$ )	
$30^{th}$ order Qcon coefficient ( $a_{13}$ )	
Number of terms to use in the expansion $(>2, <13)$ . If zero $(0)$ ,	
OpTaliX automatically determines the number of terms by searching for the	
highest order non-zero coefficient.	

Entering coefficients C1 to C32 is accomplished by the SCO command, explained in general on page 82. Specifically for Qcon surfaces the necessary commands are:

SPS QCN sij sk	Change surface profile to QCN special aspheric surface.
SCO sij sk cij coefficient(s)	Defines coefficients for SPS QCN surface(s) sij sk.

A test case, the cartesian oval, is given by Forbes [63]. This system is found in the OpTaliX examples library at  $i\$  by  $i\$  by by by  $i\$  by  $i\$  by i

Term | Qcon polynomial



Figure 8.9: Cartesian oval using Qcon parameters.

## 8.7.12 Xfreeform Asphere (SPS XFF)

The Xfreeform surface type defines a surface as combination of parts of the anamorphic (biconic) asphere, even asphere polynomials, an extended version of the XY polynomials and the Zernike standard terms. The surface sagitta is defined by:

$$z = \frac{c_{x}x^{2} + c_{y}y^{2}}{1 + \sqrt{1 - (1 + K_{x})c_{x}^{2}x^{2} - (1 + K_{y})c_{y}^{2}y^{2}}} \qquad biconic$$

$$+ \sum_{i=1}^{8} a_{i}r^{2i} \qquad even$$

$$+ \sum_{n=1}^{n \le 231} a_{n}Z_{n}(\rho,\varphi) \qquad Zernike$$

$$+ \sum_{j=0,k=0,j+k\ge 1}^{j\le 20,k\le 20} \frac{a_{jk}x^{j}y^{k}}{N^{j+k}} \qquad XY polynom$$
(8.15)

The parameters for the Xfreeform surface are defined by:

Coefficient	Definition
1	X radius = $1/c_x$
2	X conic constant = $K_x$
3	Y conic constant = $K_y$
4	$2^{nd}$ order even asphere coefficient $(a_1)$
5	$4^{th}$ order even asphere coefficient $(a_2)$
6	$6^{th}$ order even asphere coefficient ( $a_3$ )
7	$8^{th}$ order even asphere coefficient $(a_4)$
8	$10^{th}$ order even asphere coefficient ( $a_5$ )
9	$12^{th}$ order even asphere coefficient ( $a_6$ )
10	$14^{th}$ order even asphere coefficient ( $a_7$ )
11	$16^{th}$ order even asphere coefficient ( $a_8$ )
12	Zernike decenter X

continued on next page

13	Zernike decenter Y
14	Maximum Zernike terms
15	Maximum polynomial terms
16	Normalization radius
17 - 256	Zernike and polynomial terms, with Zernike terms appearing first.

The maximum number of coefficients in the Xfreeform surface is 256. Although the number of possible standard Zernike terms (max. 231) and of XY polynomials (max. 230) can be freely changed by user input in the fields no. 14 and no. 15, the sum of the Zernike and polynomial terms must obey the following condition:

 $N_{Zernike} + N_{polynom} \le 256 - 16$ 

As the Zernike terms appear first, the number of polynomial terms are limited according to the above formula.

# 8.8 Alternate Intersection Point

It is not always possible to predict the intersection point of a ray with a surface, in particular if the ray is at a high angle to the local surface axis. For example, consider the following case of a conic surface (parabola), where two intersection points are found (Fig. 8.10). Normally, the intersection point at  $P_1$  would be selected by the program which is correct. If the ray originates from 'inside' of the parabola, however, the IC command allows selecting the alternate intersection point  $P_2$  which would be more appropriate.



Figure 8.10: Selection of alternate intersection point and geometrical meaning of IC code. Left: ray starting 'outside' surface, right: ray starting 'inside' surface.

# 8.9 Axicon

Axicon surfaces are rotationally symmetric about the Z-axis and are like a cone, with the tip of the cone at the vertex of the surface. Axicons are modelled by an aspheric surface (surface type "A"). The following examples show the definition of an axicon surface by using the "EVEN" power polynomial asphere respectively the "ODD30" power ( $30^{th}$  order) polynomial asphere.

#### 8.9.1 Axicon modelled by "EVEN" Power Asphere

In the "EVEN" power polynomial asphere only the radius radius of curvature and the conic constant K need to be defined. The radius of curvature is set to a small value, the conic constant is -2 (hyperbola). As a guideline, the radius of curvature should be at least one order of magnitude smaller than the smallest radial aperture of the surface. Make sure that the radius of curvature is NOT zero!

Due to the non-zero radius of curvature there is a small deviation of the slope to that of an axicon near the tip of the cone. This deviation can be made arbitrarily small by selecting a small enough radius of curvature.

From a practical point of view, the cone angle is the most interesting parameter and the only one needed. The cone angle  $\theta$  is defined as the angle between the vertex tangent plane (i.e. the plane perpendicular to the Z-axis) and the axicon surface. This angle can be easily converted to the conic constant K by taking the limit case of the standard asphere sag (Eq. 8.1) as the radius of curvature approaches zero (curvature goes to infinity):

$$K = -\left(\frac{1}{\tan^2\theta} + 1\right) \tag{8.16}$$

Example command input:

sut s2 a	! defines aspheric surface
rdy s2 0.1	! radius of curvature should be small (but must be non-zero)
k s2 -2	! Conic constant (hyperbola)

### 8.9.2 Axicon modelled by "ODD30" Power Asphere

An alternative way of defining an axicon surface is by using the odd power special asphere (see Eq. 8.6) which accepts coefficients up to  $30^{th}$  order. Its advantage is that the tip of the axicon is exactly modelled because the ODD30 asphere also includes a linear term (slope).

sps odd s2 ! defines odd (30<sup>th</sup> order) aspheric surface

sco s2 c2 0.2 ! sets special surface coefficient C2

The cone angle  $\theta$  is related to the coefficient  $C_2$  by the relation

$$\tan(\theta) = C_2 \tag{8.17}$$

# 8.10 Hologram Surface

The optical properties of a holographic surface are based on diffraction at the effective grating spacing seen at the local intersection point of a ray. Commonly, holographic surfaces are also denoted as *diffractive* surfaces. A diffractive lens behaves like an ideal, thin refractive lens with an infinite number of focal lengths given by

$$f(\lambda) = \frac{\lambda_0 f_0}{m\lambda} \tag{8.18}$$

where  $f_0$  is the focal length at the design wavelength  $\lambda_0$  and m is the diffraction order. This result reveals the highly dispersive nature of a diffractive lens. To model these effects, several types of diffractive surfaces are available in OpTaliX.

• Linear grating (section 8.11),

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- Variable linear spacing (VLS) grating (section 8.11.1),
- Optical hologram, formed by interfering two beams of light (section 8.10.4),
- Computer-generated holograms (CGH) with a user specified radial symmetric phase distribution (section 8.10.2),
- Computer-generated holograms (CGH) with a user specified asymmetric (two-dimensional) phase distribution (section 8.10.1),
- "Sweatt" model (section 8.10.3).

Diffractive surfaces, which are represented by phase distributions  $\Phi(x, y)$ , add a phase to a ray when it strikes the diffractive surface. The direction cosines K, L, M of an impinging ray changes according to the classical grating equation, if the vectors are resolved in a rectangular coordinate system oriented with its Z-axis along the local surface normal

$$K' = K + m \cdot \frac{\lambda}{2\pi} \cdot \frac{\partial \Phi(x, y)}{\partial x}$$
(8.19)

$$L' = L + m \cdot \frac{\lambda}{2\pi} \cdot \frac{\partial \Phi(x, y)}{\partial y}$$
(8.20)

$$M' = \sqrt{1 - (K'^2 + L'^2)} \tag{8.21}$$

where  $\lambda$  is the wavelength and m is the diffraction order. The partial derivatives of the function  $\Phi(x, y)$  are proportional to the local grating frequencies  $\nu_x, \nu_y$ 

$$\nu_x = \frac{\Phi(x, y)}{x}, \qquad \nu_y = \frac{\Phi(x, y)}{y} \tag{8.22}$$

and we have

$$K' = K + m \cdot \frac{\lambda}{2\pi} \cdot \nu_x \tag{8.23}$$

$$L' = L + m \cdot \frac{\lambda}{2\pi} \cdot \nu_y \tag{8.24}$$

Note, that the phase function  $\Phi$  is expressed in terms of the **absolute** optical path difference (OPD), i.e. in lens units. A more detailed treatment of vector ray tracing through general holograms is given by Welford [58].

Some other programs define the phase in units of the reference/design wavelength. For such cases the hologram coefficients must be normalized to the design wavelength first before they can be used in OpTaliX. This is accomplished by the relation

$$c_i(OpTaliX) = \frac{c_i(other)}{\lambda_0} = \frac{c_i(other)}{HWL}$$
(8.25)

with  $\lambda_0 = HWL$  given in  $\mu m$ .

Note also that diffractive structures (holograms, grating, etc.) exhibit a significant variation of diffracted energy depending on wavelength, incidence/diffraction angle, diffraction order and on the

grating structure. This effect is accounted for in transmission analysis (page 335). A detailed description of the relevant theory is given in sect. 8.11.3 (page 95).

### **Hologram Data Entry:**

The nomenclature for hologram surfaces is uniform throughout all types of holograms, including linear (straight-line ruled) gratings.

HCO sij cij coeff	Hologram coefficients cij on surface(s) sij
	Alternative form of entering HOE-coefficients, where "i" denotes
	a coefficient number. For example, HC12 is coefficient no. 12.
	This form is particularly useful for defining coefficients as vari-
HCi sij coeff	ables in optimization.
	The following commands are synonymous :
	HC7 s4 0.1234e-3
	HCO s4 c7 0.1234e-3
	Hologram type, designating which phase function is used.
	htype = $0$ : linear grating, see section 8.11,
	htype = 1: symmetrical phase function as defined in Eq. 8.26,
	htype = 2 : asymmetrical (2d) phase function as defined in sec-
HOI [SI]] htype	tion 8.10.1.
	htype = 3 : two-point hologram defined by object and reference
	point source.
	htype = 4 : VLS-grating (see section 8.11.1).
HWL sk design_wavel	Hologram design wavelength at surface sk, in micrometers.
HOR [sk sij] order	Hologram order, an integer value. Note that the sign of the
	hologram order must be changed if the orientation of the HOE
	changes between setups and the local surface normal points in
	the opposite sense.
GRO [sk sij] order	Creting order or interconvolue. This commond is sheelets but
	Grating order, an integer value. This command is obsolete, but
	still available. Use HOR instead.
GRX [SK S1]]	Grooves per mm, the diffraction is seen in the X-direction.
GDV [ablainin]	
GRI [SK SI]]	Grooves per mm, the diffraction is seen in the Y-direction.
grooves_per_hun_r	V coordinate of chiest point source for helegraphic surface
HXI SI J ODJ_SOURCE_X	A-cooldinate of object point source for holographic surface.
	of the hologram surface
UV1 ci i obi cource u	V goordingta of object point source for belographic surface.
hii sij obj_source_y	ability of object point source for horographic surface.
	tem of the hologram surface
	Z coordinate of object point source for holographic surface
1121 SIJ ODJ_SOULCE_Z	abj source w is given relative to the local coordinate swa
	tem of the hologram surface
UV2 ci i rof course u	V coordinate of reference point source for holographic surface
nAZ SIJ LELSOULCE_X	x-coordinate of reference point source for holographic surface.
	of the hologram surface
	of the hologialli sufface.
1	continued on next page

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HY2 sij ref_source_y	Y-coordinate of reference point source for holographic surface.
	ref_source_y is given relative to the local coordinate system
	of the hologram surface.
HZ2 sij ref_source_z	Y-coordinate of reference point source for holographic surface.
	ref_source_y is given relative to the local coordinate system
	of the hologram surface.
HV1 sij rea vir	Defines object point course of real (DEA diverging beem) or
	virtual (VID, converging beem) for the designated surface(a)
	virtual (virk, converging beam) for the designated surface(s).
	Defines reference point source as real (REA, diverging beam)
	or virtual (VIR, converging beam) for the designated surface(s).
SUT [sij] SG	Set surface type to put a grating on a (spherical) base surface
	as given in the example command to the left. See also the full
	description of the SUT command, page 65.
SUT [sij] SH	Set surface type to put a general hologram (including grating)
	on a spherical base surface as given in the example command
	to the left. See also the full description of the SUT command,
	page 65.
BLD [sk sij] depth	
	Blaze depth in mm. Required in transmission/efficiency calcu-
	Blaze type used for diffraction efficiency calculations. Specifies
	the diffractive structure as
	IDL : 100% of the diffracted energy is directed into the specified
BLT [sk s1]	grating order (GRO/HOR) at all wavelengths.
[IDL KIN STE SIN]	KIN : Kinoform (sawtooth) profile,
	STE : step approximation of the Kinoform profile,
	SIN : sinusoidal profile.
BLN [sk sij] levels	Number of discrete levels in the step approximation of a Kino-
	form diffracting profile
HPH [sk si. i]	
	Plot hologram phase.
HPHN sj xabs yabs	
	Returns the phase (in waves) on a diffractive/holographic sur-
	tace sj
HZO [sk sij]	Calculate zones in radial holograms
VLS [sij] c 3 c 4	Adds properties of a variable linear spacing (VLS) grating to
c_10	a surface, i.e. converts a surface to a VLS grating. Surface
	type and hologram type are automatically set and do not require
	any further user interaction. The coefficients $c_3$ to $c_10$ are
	defined in Eqs. 8.34 and 8.35 respectively. For example, c_3
	defined in Eqs. 8.34 and 8.35 respectively. For example, c_3 defines the constant grating frequency in grooves/mm.

#### 8.10.1 Asymmetric Phase Function

The function for a generally asymmetric phase is defined by a polynomial function of up to 28 coefficients:

$$\begin{split} \Phi(x,y) &= & a_1 \\ & & a_2x + a_3y \\ & & a_4x^2 + a_5xy + a_6y^2 \\ & & a_7x^3 + a_8x^2y + a_9xy^2 + a_{10}y^3 \\ & & a_{11}x^4 + a_{12}x^3y + a_{13}x^2y^2 + a_{14}xy^3 + a_{15}y^4 \\ & & a_{16}x^5 + a_{17}x^4y + a_{18}x^3y^2 + a_{19}x^2y^3 + a_{20}xy^4 + a_{21}y^5 \\ & & a_{22}x^6 + a_{23}x^5y + a_{24}x^4y^2 + a_{25}x^3y^3 + a_{26}x^2y^4 + a_{27}xy^5 + a_{28}y^6 \end{split}$$

Note that the phase is a function of x and y and not z, and thus is independent of the substrate shape. Individual coefficients  $a_i$  are entered by the commands HCi or HOC (see also section 8.10 for a complete description of the commands).

Also note that the phase is defined in absolute (lens) units (i.e. typically in mm).

#### **Example:**

sut	s2	SH	! base surface is spherical with superimposed hologram
HC3	s1	0.123	! Hologram coefficient c3 ( $a_3$ term) on surface 1 is 0.123
HOC	s1	c3 0.123	! As above

#### 8.10.2 Symmetric Phase Function

The phase function of a symmetric hologram takes the absolute value of a power series expansion in the radial coordinate h.

$$\Phi(x,y) = a_1 + a_2h + a_3h^2 + a_4h^3 + a_5h^4 + a_6h^5 + \dots$$
(8.26)

where  $h = \sqrt{x^2 + y^2}$ 

In the paraxial domain the properties of a lens are completely described by the  $a_3$  term and the diffractive lens power  $\varphi_{diff}$  is given by

$$\varphi_{diff} = \frac{1}{f} = -2ma_3\lambda \tag{8.27}$$

where m is the diffraction order.

The blaze depth d, i.e. the sagitta of the radial groove profile, is then calculated by [62],

$$d = \frac{\lambda_0}{n_0 - 1} \tag{8.28}$$

where  $\lambda_0$  is the reference wavelength, and  $n_0$  is the refractive index at the reference wavelength. See also sect. 23.3 about manufacturing aspects and calculation of diffraction zones related to diffractive structures. This section also describes conversion of hologram coefficients to other programs.

#### 8.10.3 Sweatt Model

An alternative to the phase models described in the previous sections is to using the so-called *Sweatt model*. It has been shown by Sweatt [52, 53] and Kleinhans [26] that a diffractive lens is mathematically equivalent to a thin refractive lens, provided the index of refraction goes to infinity. For practical

cases a very high refractive index (n = 10000) is used. This reduces the lens thickness profile and introduces an appreciable shape over a relatively small physical path length. The advantage of this method is, that it allows the use of existing ray tracing routines for designing diffractive lenses. The chromatic properties of the diffractive lens are modelled by

$$n_s(\lambda, m) = m \frac{\lambda}{\lambda_0} \left[ n_s(\lambda_0) - 1 \right] + 1$$
(8.29)

where the subscript s refers to the "Sweatt" model and  $\lambda_0$  is the design wavelength. The refractive index is proportional to the wavelength. It is implicitly assumed that the design order is the first order. The lens curvatures of the equivalent "Sweatt" model for a given lens power  $\varphi$  at the design wavelength are given by

$$c_{1,2} = c_s \pm \frac{\varphi_0}{2 \left[ n_s(\lambda_0) - 1 \right]}$$
(8.30)

where  $c_s$  is the curvature of the diffractive substrate. Higher order terms in the diffractive surface phase polynomial are modelled by aspherization of the base surface.

To simplify the set up of the "Sweatt" model, a material (glass) SWEATT is available. Enter gla sk sweatt in the command line to convert a surface sk to the "Sweatt" model. Alternatively, enter the material (glass) name in the appropriate row/column of the surface spreadsheet editor.

#### Example:

sut	s2	S	! Base surface is spherical. Note, that the surface type "H" is not
			required in the Sweatt model
gla	s2	sweatt	! Defines the high-index glass "SWEATT"
hwl	s2	0.633	! Design wavelength used in the Sweatt model is 0.633 $\mu m$

### 8.10.4 Two-Point Hologram

This type of holographic surface describes the interference pattern of two point sources, i.e. two spherical waves, which includes plane wavefronts as the limiting case. The local grating frequency is determined by the location and orientation of the resultant interference fringes. To model a two-point hologram, the location of the two sources and the wavelength of the source beams must be given. The sources used to record the hologram are specified by X-, Y- and Z-coordinates relative to the local coordinate system of the holographic surface. The parameters are HX1, HY1, HZ1 for the object point source and HX2, HY2, HZ2 for the reference point source.

The parameters HV1 and HV2 define from which side each beam is directed during construction. Point sources are considered *real* if the beam is diverging from the source, or *virtual* if the beam is converging toward the source.

Tracing a ray through a holographic surface makes use of the information about the geometry of formation of the hologram. Unlike to phase models, the local fringe spacing is not explicitly computed . Holograms can be applied to surfaces of any arbitrary shape.

We follow the notation by Welford [58] and let n be a unit vector along the local normal to the hologram surface (see Fig. 8.11). The hologram is recorded by two spherical wavefronts emerging from the object point source and the reference point source, represented by the vectors  $r_o$  and  $r_r$ . The unit vectors  $r'_o$  and  $r'_r$  represent the reconstruction and image rays at the intersection point P. The image ray  $r'_r$  is obtained by the equation

$$n \times \left(r'_o - r'_r\right) = \frac{m\lambda'}{\lambda} n \times (r_o - r_r) \tag{8.31}$$

where m is the order of diffraction,  $\lambda$  is the recording wavelength (design wavelength HWL) and  $\lambda'$  is the reconstruction wavelength.

In a coordinate system oriented with its Z-axis to the local surface normal at P the vectors are resolved into two components

$$K'_0 - K'_r = \frac{m\lambda'}{\lambda}(K_0 - K_r)$$
 (8.32)

$$L'_0 - L'_r = \frac{m\lambda'}{\lambda}(L_0 - L_r)$$
 (8.33)

of a typical unit vector (K,L,M).



Figure 8.11: Notation for ray tracing at a holographic surface.

### Example using a two-point model:

sut s2 SH	! base surface is spherical with superimposed hologram
hot s2 3	! Hologram type specifies "two-point" hologram
hz1 s2 -1.e20	! Object point source is at infinity, object wavefront is flat.
hz2 s2 50	! Reference point source is at +50 mm with respect to surface vertex.
hvl rea	! Real object point source.
hv2 rea	! Real reference point source.
T ( ) ( ) ( )	

Note, that all other point source parameters (HX1,HY1, HX2,HY2) are initially zero.

### **Design Example:**

An example holographic lens is found in the directory <code>\$i\examples\diffractive\two-point-hoe.otx</code>.

The diffractive optical element (DOE) is recorded with a He-Ne laser at a wavelength  $0.6328\mu m$ . The location of the point sources are specified in the local coordinate system of the holographic optical element (HOE).

We also note the hologram construction parameters as shown in the surface listing (see LIS command):

```
# Hologram coefficients :

1 HOT 3 HOR -1 HWL 0.63300

HX1 0.0000 HX2 0.0000

HY1 0.0000 HY2 0.0000

HZ1 -0.10000E+21 HZ2 50.000

HV1 REA HV2 REA
```



Figure 8.12: Two-point hologram on curved substrate. See example file at \$i\examples\diffractive\two-point-hoe.otx

Since this is an on-axis lens, the location of the point sources of the recording laser beams are at HX1 = HY1 = 0, and HX2 = HY2 = 0. Point source 1 is at infinity ( $HZ1 \ 0$ ), so it is actually a plane wave at the hologram surface. Point source 2 is located at the focal point, which is 50mm to the right of the HOE ( $HZ2 \ 50.0$ ). Based on elementary holography theory, the plane wave incident to the hologram will be diffracted into a spherical (on-axis) wave converging to the focal point and thus constructing a perfect image.

We also note the curvature of the hologram surface. For on-axis imaging it does not make any difference whether the hologram surface is curved or not, since the hologram is recorded by two (perfect) point sources located on the axis. In this case the reconstruction geometry is identical to the recording geometry. For off-axis imaging, however, a curved hologram substrate is analogous to "bending" of a thin lens and yields coma-free and aplanatic imaging.

# 8.11 Diffraction Grating Surface

Diffraction gratings are a subset of holographic surfaces and are used to model straight-line ruled gratings. This simplifies data entry without the need to fully specify complex holograms. However, gratings may also be specified by an asymmetric hologram surface (see section 8.10.1, in which the linear coefficients *a*2, *a*3 directly give the grating frequency in X- and Y-direction. The straight rules may have any orientation with respect to the base surface (respectively the local coordinate system). The orientation is defined by proper setting of the grating frequency in X- and Y-direction (GRX, GRY). The grating frequency is always defined on the surface tangent plane in lines (grooves) per

millimeter.

GRX	[sij]	grooves_per_mm_X	Grooves per mm, the diffraction is seen in the X-direction.
GRY	[sij]	grooves_per_mm_Y	Grooves per mm, the diffraction is seen in the Y-direction.
HOR	[sij]	order	Hologram diffraction order, an integer value.
SUT	[sij]	SG	Set surface type to put a grating on a (spherical) base surface as given in the example command to the left. See also the full description of SUT command (page 68).

### Example:

sut	s2	SG	! base surface is spherical with grating additive
hor	s2	1	! Diffraction order is +1
gry	s2	100	! Grating frequency is seen in Y-direction at 100 Lines/mm.
grx	s2	55	! Grating frequency is seen in X-direction at 55 Lines/mm.

## 8.11.1 Variable Line Spacing (VLS) Grating Surface

A linear variable spacing grating (VLS-grating) is a special form of a straight-line ruled grating (see previous section). The phase is described by a polynomial function

$$\Phi(y) = a_3y + a_4y^2 + a_5y^3 + a_6y^4 + a_7y^5 + a_8y^6 + a_9y^7 + a_{10}y^8$$
(8.34)

The grating frequency  $\nu_y$  is the first derivative of  $\Phi$ 

$$\nu_y = a_3 + 2a_4y + 3a_5y^2 + 4a_6y^3 + 5a_7y^4 + 6a_8y^5 + 7a_9y^6 + 8a_{10}y^7$$
(8.35)

Note that a VLS-grating is only defined in the Y-direction. Arbitrary orientations of the grooves can be simulated by applying a Z-rotation to the surface (see CDE command). Also note that the coefficients numbering starts at 3, which ensures consistency with the definitions of the conventional grating (sect. 8.11) and the asymmetric phase function (sect. 8.10.1).

The grating frequency  $\nu_y$  is always defined on the tangent plane of a surface. If only  $a_3$  is specified, the VLS-grating behaves like a straight-line ruled gratings with constant groove spacing (grating frequency =  $a_3$  in grooves/mm).

A VLS-grating is traced in OpTaliX similarly to an asymmetric phase hologram. Therefore the surface type must be "H".

Example:

sut	s2	SH	! base surface is spherical plus hologram
hor	s2	1	! Diffraction order is +1
hot	s2	4	! Hologram type is VLS-grating
hco	s2	c3 100	! Hologram coefficient 3 (equivalent to the grating frequency = 100 grooves/mm).
hc3	s2	100	! as above.

A simplified form of entering/defining VLS gratings is provided by the following command:

VLS [sij] c_3 c_4 Ac c_10 gr gr ica tic 8	adds properties of a variable linear spacing (VLS) rating to a surface, i.e. converts a surface to a VLS rating. Surface type and hologram type are automat- cally set and do not require any further user interaction. The coefficients $c_3$ to $c_10$ are defined in Eqs34 and 8.35 respectively. For example, $c_3$ defines the constant grating frequency in grooves/mm
----------------------------------------------------------	---------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------

#### 8.11.2 Conversion of Coefficients for a VLS Grating

A different form of describing VLS-gratings on a curved substrate is occasionally used. It is given by Kita et.al. [25]

$$\sigma = \frac{\sigma_0}{\left(1 + \frac{2b_2w}{R} + \frac{3b_3w^2}{R^2} + \frac{4b_4w^3}{R^3}\right)}$$
(8.36)

where the groove spacing  $\sigma$  is defined as a function of the local coordinate w measured from the center of the grating and the radius of curvature R of the concave grating surface. The coefficients  $b_2, b_3, b_4$  are easily converted to the form used in OpTaliX (Eq. 8.35)

In the Kita paper, the groove spacing  $\sigma$  is defined as a function of the local coordinate w measured from the center of the grating and the radius of curvature R of the concave grating surface, whereas in OpTaliX the groove spacing is expressed by the grating frequency  $\nu$ 

$$\nu_y = a_3 + 2a_4y + 3a_5y^2 + 4a_6y^3 + \dots \tag{8.37}$$

Groove spacing and (local) grating frequency are related by  $\nu = 1/\sigma$ . Inserting into Eq. 8.36 and rearranging yields

$$\nu = \nu_0 + \frac{2\nu_0 b_2}{R}y + \frac{3\nu_0 b_3}{R^2}y^2 + \frac{4\nu_0 b_4}{R^3}y^3$$
(8.38)

A deeper analysis indicates that the conventions of the coordinate axes used in the paper by Kita and those used in OpTaliX are different. Obviously w = -y. Thus, we modify Eq. 8.38 accordingly

$$\nu = \nu_0 - \frac{2\nu_0 b_2}{R}y + \frac{3\nu_0 b_3}{R^2}y^2 - \frac{4\nu_0 b_4}{R^3}y^3$$
(8.39)

Comparing Eqs. 8.35 and 8.39, the conversion formulas are directly obtained as

$$a_{3} = \nu_{0} = 1/\sigma_{0}$$

$$a_{4} = -\frac{\nu_{0}b_{2}}{R} = -\frac{b_{2}}{\sigma_{0}R}$$

$$a_{5} = \frac{\nu_{0}b_{3}}{R^{2}} = \frac{b_{3}}{\sigma_{0}R^{2}}$$

$$a_{6} = -\frac{\nu_{0}b_{4}}{R^{3}} = -\frac{b_{4}}{\sigma_{0}R^{3}}$$
(8.40)

#### **Numerical Example:**

We use the data given in the paper by Kita 8.36: R = 5649mm,  $\sigma_0 = 1/1200mm$ ,  $b_2 = -20$ ,  $b_3 = 4.558 \cdot 10^2$ ,  $b_4 = -1.184 \cdot 10^4$ . The following table shows the analytically converted coefficients.

OpTaliX	calculated
Coeff.	from Eq. 8.40
$a_3$	1200
$a_4$	4.2485
$a_5$	$1.714 \cdot 10^{-2}$
$a_6$	$7.882 \cdot 10^{-5}$

### 8.11.3 Diffraction Efficiency Calculation

OpTaliX calculates the *scalar* diffraction efficiency on surfaces that contain diffractive structures (hologram, grating). Diffraction efficiency describes the amount of energy associated to a ray when passing a diffractive structure. Diffraction efficiency depends on wavelength, incidence angle, diffraction order and on the profile of the diffractive structure. The scalar model implemented in OpTaliX currently does not include variations due to polarization state.

The results of diffraction efficiency calculations are included in transmission analyses (requires settings TRA Y and POL Y).

The following profiles of diffractive structures are currently available:

- Sawtooth Profile (Kinoform Blaze Type)
- Sawtooth Step Approximation
- Sinusoidal Profile

### 8.11.3.1 Sawtooth Profile (Kinoform)

The diffraction efficiency into the  $m^{th}$  diffracted order of a sawtooth (Kinoform) profile (Fig. 8.13) is approximated by

$$\eta(m) = \left(\frac{\sin\left[\pi(\alpha - m)\right]}{\pi(\alpha - m)}\right)^2 \tag{8.41}$$

with:

 $\alpha$ 

 $= \frac{d_1 \left( n_1 \cdot \cos\theta_1 - n_2 \cdot \cos\theta_2 \right)}{\lambda}$ 

$$m = \text{diffracted order (GRO or HOR)}$$

 $d_1$  = blaze depth (BLD)

 $n_1$  = refractive index before surface

 $n_2$  = refractive index after surface

 $\lambda$  = wavelength

- $\theta_1$  = local incidence angle of ray
- $\theta_2$  = local diffraction angle of ray

Within each period, the profile is a linear function of the spatial coordinate x. The blaze depth  $d_1$  (BLD command) of the local grating structure is always measured to the local surface normal.



Figure 8.13: Sawtooth profile of a diffracting structure (Kinoform structure)

#### 8.11.3.2 Sinusoidal Profile

The diffraction efficiency into the  $m^{th}$  diffracted order of a sinusoidal profile (Fig. 8.14) is approximated by

$$\eta(m) = [J_m(\pi \cdot \alpha)]^2 \tag{8.42}$$

where  $\alpha = \frac{d_1 \left( n_1 \cdot \cos \theta_1 - n_2 \cdot \cos \theta_2 \right)}{\lambda}$ , and  $J_m$  is the Bessel function of first kind, order m.



Figure 8.14: Sinusoidal profile of a diffracting structure.

#### 8.11.3.3 Step Approximation

The step approximation of a Kinoform profile is specified by the BLT STE command. The diffraction efficiency into the  $m^{th}$  diffracted order of a step approximation of a Kinoform profile (Fig. 8.15) is approximated by

$$\eta(m) = \left[\frac{\sin(m\pi/N)}{m\pi}\right]^2 \cdot \left[\frac{\sin(\pi(\alpha-m))}{\sin(\pi(\alpha-m)/N)}\right]^2$$
(8.43)

where:

N = number of discrete levels in each grating period (BLN command).

$$\alpha = \frac{d_1 \left( n_1 \cdot \cos\theta_1 - n_2 \cdot \cos\theta_2 \right)}{\lambda}$$

- m = diffracted order (commands GRO or HOR)
- $d_1$  = blaze depth (BLD command)
- $n_1$  = refractive index before surface
- $n_2$  = refractive index after surface
- $\lambda$  = wavelength
- $\theta_1$  = local incidence angle of ray
- $\theta_2$  = local diffraction angle of ray



Figure 8.15: Step approximation profile of a Kinoform diffracting structure.

### 8.11.3.4 Diffraction Efficiency Example

The effect of diffraction efficiency at diffractive structures (hologram, grating, etc.) can be best demonstrated with transmission analysis vs. wavelength. Load the example file

\$i\examples\spectrometer\rowland-grating.otx.

The optical system, as shown in Fig. 8.16 contains a linear grating on a curved surface. The necessary parameters required to analyze diffraction efficiency effects are blaze type (BLT) and blaze depth (BLD):

BLT s1 KINBlaze type is KinoformBLD s1 0.00027Blaze depth is 0.00027 mm

Transmission analysis vs. wavelength is then accomplished by the command:

TRA LAM

See Fig. 8.17 for the corresponding transmission curve.

# 8.12 Fresnel Surface

In a Fresnel lens the curved surface of a lens is collapsed in annular zones to a thin plate. As shown in Fig. 8.18, this has the refracting effect of the lens without its thickness or weight. Such lenses are often used as condensors in overhead projectors, spotlights and signal lamps.

A Fresnel lens is defined by the radius of curvature R of the refracting surface (as it would be defined for a conventional lens) and the depth d of the annular zones (see Fig. 8.18).

FTH fresnel_depth	Fresnel thickness, that is the depth or thickness of the annular rings.
	Smaller values for FTH result in a finer radial spacing of the annular
	zones. This option is currently only available in the command line. It
	cannot be set from the menu. Note that the surface type (SUT) must
	be "F" in conjunction with the "S" or "A" qualifier for the surface
	shape ( $S =$ spherical, $A =$ aspherical).



Figure 8.16: Rowland grating.

Note, that "shadowing" effects due to the finite thickness of the structure are not taken into account during ray tracing.

#### **Example input:**

sut	s1	SF	! defines a Fresnel surface with spherical base curvature
rdy	s1	30	! defines base radius, which controls refraction
fth	s1	1	! depth of annular zones

# 8.13 Total Internal Reflection (TIR) Surface

Total internal reflection (TIR) occurs on glass-air interfaces when the angle of incidence in the medium of higher index exceeds the critical angle  $\theta_c$ . Under that condition there can be no refracted light and every ray undergoes total reflection as shown in Fig. 8.19.

The critical angle is calculated by

$$\sin(\theta_c) = \frac{n}{n'} \tag{8.44}$$

A TIR surface always behaves like a mirror surface, except that TIR condition is calculated to determine whether a ray is valid or is blocked. Thus, rays that hurt the TIR condition (i.e. the angle of incidence is less than  $\theta_c$  are blocked whereas rays at  $\theta > \theta_c$  is reflected.

A TIR surface is defined by the following command:



Figure 8.17: Diffraction efficiency calculation on a Rowland grating with a "Kinoform" profile.

TIR sk sij or RMD TIR sk sij	Defines total internal reflecting surface (TIR). Adds "T" to surface type. A TIR surface behaves like a mirror surface except that rays only pass if TIR condition is fulfilled. See also RMD TIR, respectively REFL and REFR to convert a surface to reflecting or refracting mode. Calculating TIR condition requires proper definition of both materials, GL1 and GL2, where, according to Eq. 8.44, $n =$ index of GL1 and n' = index of GL2. By default, $n' = 1$ .
	The TIR flag is ignored at non-sequential surfaces as the TIR condition is <i>always</i> checked and the corresponding ray direction is automatically chosen.

Light is totally reflected, i.e. R = 1, if the TIR condition according to Eq. 8.44 is fulfilled, however, there is a phase change on reflection which depends on incidence angle, wavelength and which is different for S- and P-components (polarized light). The phase changes are calculated by [4]

$$\tan\frac{\delta_1}{2} = -\frac{\sqrt{\sin^2\theta_i - n^2}}{n^2 \cos\theta_i} \tag{8.45}$$

$$\tan\frac{\delta_2}{2} = -\frac{\sqrt{\sin^2\theta_i - n^2}}{\cos\theta_i} \tag{8.46}$$

where the subscript (1) means S-polarization (German: *senkrecht*) and (2) means P-polarization (German: *parallel*).

Although there is no loss of light at TIR, the wavefront (i.e. phase) is altered according to Eqs. 8.45 and 8.46. For unpolarized light, the impact on wavefront  $\Delta w$  is given by

$$\Delta w = \frac{\left(\delta_1 - \delta_2\right)\lambda}{2\pi} \tag{8.47}$$



Figure 8.18: Fresnel lens and construction method of annular zones.



Figure 8.19: Total internal reflection (TIR) condition.

The phase change is **always** applied, irrespectively of whether polarization ray trace is enabled or not (see POL).

An example showing the effect on wavefront is provided in *\$i\examples\misc\tir.otx*. The results are shown in Fig. 8.20

Even though the aspheric lens should provide a near perfect image, the coma-like tail appearing on the PSF in Fig. 8.20 is caused by wavefront (phase) variation as a function of incidence angle variation across the pupil, in particular by those rays striking the TIR surface in the neighborhood of the critical angle  $\theta_c$ . Note that the focussed spot of Fig. 8.20 is not centered on the optical axis but is shifted. This shift is known as the Goos-Hanchen effect. Similarly, we may explain this effect in the language of Fourier-Transform theory by multiplying a function (the wavefront) by a linear phase factor. See also Mansuripur [36] for a more thorough explanation of this effect.

# 8.14 Non-Sequential Surface

Non sequential surfaces (NSS) are a special subset of the total lens, where the sequence of the surfaces, which are hit by a ray, is determined by the light ray itself. This means that the program automatically determines which surface is hit next.

Command Overview:



Figure 8.20: Total internal reflection example. See *\$i\examples\misc\tir.otx*. Shows optical layout (left), wavefront (right) and point spread function (underneath).

OpTaliX

NSS sij	Converts a group of (previously entered) sequential surfaces
	into an equivalent NSS-range. The command automatically
	sets the correct tilt types on entrance port and exit port. The
	non-sequential surface range may also include the object sur-
	face (e.g. NSS s08), however, ray aiming is unlikely to
	work properly in this case. The NSS s0k option is mainly
	useful in illumination applications with predefined rays (see
	also source rays, page 311).
DEL NSS sij	Converts a group of non-sequential surfaces into sequential sur-
	faces. Tilts and decenters are appropriately changed to reflect
	the sequential model. If there is more than one NSS range in an
	optical system, each range must be separately converted. Thus,
	it is not allowed to convert the whole surface range spanning
	the NSS sub-ranges.
GL1 sij glass-name	Define glass on the "left side" (i.e. the side with negative local
	Z-axis) of the surfaces sij
GL2 sij gl-name	Define glass on the "right side" (i.e. the side with positive local
	Z-axis) of the surfaces sij
MXH sij max_hits	Maximum number of hits allowed for each surface in a NSS- range before declaring a ray failure. Note that each non- sequential surface may be assigned a different value for MXH. Ray tracing may also be terminated if a surface with absorbing (obstructing) property is hit.

Add "N" to the surface type (SUT) to specify a non-sequential surface. In OpTaliX non-sequential surfaces are always handled as decentered surfaces, even where all decenter/tilt data on a designated surface are zero. Thus, the surface type qualifier "D" must always be specified in conjunction with non-sequential surfaces. Consecutive non-sequential surfaces are defined in a NSS-range. The number of NSS-ranges within an optical system is unlimited. Fig. 8.21 shows the definition of non-sequential surface and an exit port surface. The entrance port surface is sequential, since it is the last surface of the sequential range. The exit port surface is non-sequential, since it is the last surface of the NSS-range. All surfaces entered between the entrance- and exit- port surface are non-sequential. Within a specified NSS-range, they may be entered in any order and may be arbitrarily tilted and decentered. The entrance port and exit port surfaces must have the tilt mode NAX, whereas for all other surfaces within a NSS-range the tilt mode DAR must be selected. NAX and BEN tilt modes are not allowed in a NSS-range!

## 8.14.1 Converting Sequential Surfaces to Non-sequential Surfaces

A range of sequential surfaces is converted to non-sequential surfaces by the command NSS si...j. This conversion automatically performs the following steps:

- set the glasses GL1 and GL2,
- set the tilt modes (TLM) of all surfaces inside the NSS-range to DAR,
- set the tilt modes (TLM) of entrance port and exit port to NAX,
- freezes all apertures (i.e. all apertures of surfaces inside the NSS-range are checked if a ray hits the surface inside the aperture (valid) or outside (invalid),

• refer all non-sequential surface vertex coordinates locally to the entrance port.

Also note that all surfaces in the range must be sequential surfaces. Ranges containing both sequential and non-sequential surfaces (before conversion is attempted) may lead to unexpected results, because they cannot be unambiguously converted.

# 8.14.2 Non-Sequential Coordinate System

The entrance port surface defines a new (local) coordinate system for all subsequent surfaces within a NSS-range. The origin is at the vertex of the entrance port surface. All non-sequential surfaces in a given NSS-range are entered by specifying their X, Y and Z decenters (XDE,YDE,ZDE) and their Euler rotation angles (ADE,BDE,CDE) with respect to this (local) coordinate system. Note that the separation (THI - command) has no meaning for NSS and is (must) therefore set to zero for all non-sequential surfaces. The THI-values are ignored within a NSS range. To specify the Z-location of a non-sequential surface relative to the entrance port coordinate system, use the ZDE command instead.

The exit port surface, being of type non-sequential, defines a new coordinate system for the following sequential surfaces. The origin is at the vertex of the exit port surface. The entrance port surface and the exit port surface must not be mirror surfaces. The image surface must be sequential. NSS-ranges must not overlap.



Figure 8.21: Definition of non-sequential surface range.

# 8.14.3 Glass Specification for Non-Sequential Surfaces

With a NSS-range, two glasses must be specified for each non sequential surface: The GL1 command specifies the glass on the "left side" of the surfaces (the side containing the negative local Z-axis). GL2 specifies the glass for the opposite side (positive local Z-axis).

# 8.14.4 Transfer between Non-Sequential Surfaces

At a given surface, the program traces the intersection points of a ray with all other surfaces within a NSS-range. On the basis of this information, the transfer of a ray from one NSS to the next NSS is determined by the following criteria:

The optical path difference (OPD) must always be positive. "Virtual" ray trace within a NSS-range is not allowed. If more than one surface with positive OPD exist, the surface with the smallest OPD

is selected. It is not possible to ignore aperture violations (i.e. a ray falls outside of the valid aperture definition). The ray intersection point must always be within the valid aperture definition. A ray can hit the same surface two or more times in succession without having to transfer to another surface.

Entrance port surface :	The surface is always a sequential surface (since it is the last surface of the sequential range) and of type "SD" or "AD". It defines a new axis and a new origin for all subsequent surfaces in the NSS-range. The tilt modus (TLM) is 1 (NAX), defining a new coordi- nate system, with its origin at the vertex of the en- trance port surface.
Exit port surface :	The surface is always a non-sequential surface (since it is the last surface in the NSS-range) and decentered. ( $TLM = 1$ ).
All other surfaces in NSS-range :	Surfaces are always referred to the origin (local ver- tex coordinates) of the entrance port surface.

# 8.14.5 Absorbing (obstructing) Surface Property

An absorbing property may be assigned to a non-sequential surface by declaring the primary aperture (pupil) p1 on a surface obstructing. For example,

cir s3 obs

sets the aperture type (property) of a circular aperture to obstructing. A ray which hits an absorbing (obstructing) surface is terminated on that surface.

## 8.14.6 General Notes on Non-Sequential Ray Tracing

The object surface and the image surface cannot be included in a non-sequential range.

It is possible to set up non-sequential ranges such that a ray that enters cannot exit. To avoid infinite ray trace loops, a maximum of hits on a given surface can be specified. See the MXH command, which provides a means to terminate non-sequential ray tracing after a certain number of surface hits.

Pupil finding may be unpredictable whenever the stop is a non-sequential surface or follows a non-sequential surface. It is recommended that the stop is placed ahead of any non-sequential range whenever possible.

# 8.15 Pickup Surfaces

The parameters of a surface can be made dependent on the setting of another surface. This is particularly useful in double pass or symmetrical systems where surface parameters, such as curvature, thickness, tilt/decenter, material, aspheric coefficients, are specified by a linear relationship with parameters on a preceding surface. In the simplest case, the value of a parameter can be directly copied (picked up) from another (preceding) surface, however, its value may also be negated or scaled by a factor.

A pickup is used to specify a particular surface parameter (such as a radius) by the value of another surface parameter of the same kind (e.g. another radius). The parameter to be picked up is an *independent* parameter, as its value can be independently specified. The parameter defined at the pickup

surface is the *dependent* parameter as its value is permanently updated on changes of the independent parameter.

Pickups can be applied to a group of surface parameters, for example to all tilt/decenters (XDE, YDE, ZDE, ADE, BDE, CDE) as a whole, or may be individually specified for single parameters (for example XDE only).

Surface pickups are specified by the commands:

	Pickup parameter XXX for surface sk from surface sj. Op- tional parameter:
PIK XXX sk sj [ A [ B ]] or	A: Multiply by value A (default 1.0) B: Add offset B (default 0.0) DEC: Pickup all decenter data as a group
PIK DEC sk sj [A]	ASP: Pickup all aspheric coefficients as a group.
or	Examples:
PIK ASP sk sj	PIK THI s4 s3 PIK CUY s4 s3 -1.0 PIK GLA s4 s3
LIS PIK [sk sij]	
or PKL	List pickups.
DEL PIK XXX [sk sij]	Delete all pickups denoted by XXX parameter in the specified surface range.

### Notes:

- If the dependent surface is not already decentered, it is automatically converted to a decentered surface (i.e. adds the "D" qualifier to the surface type, see sect. 8.6).
- If the dependent surface is not already an aspheric surface, it is automatically converted to an aspheric surface (i.e. adds the "A" qualifier to the surface type, see sect. 8.6).

Pickups may be entered in any order and pickups can be chained. That is, a dependent parameter can become the independent parameter of an other pickup. For example, the independent pickups

PIK CUY s3 s1 PIK CUY s5 s1

are equivalent to chaining pickups

PIK CUY s3 s1 PIK CUY s5 s3

Pickups may also be defined in reverse order. For example,

PIK THI s3 s4

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Circular pickups are not allowed. For example,

PIK CUY s3 s2 PIK CUY s2 s3

#### More Examples:

PIK CUY	s5 s4	The curvature of surface 5 is picked up from surface 4.
PIK THI	s3 s2 -1.0	The distance of surface 3 is picked up from surface 2 with opposite sign of surface 2.
PIK ASP	s3 s1	All aspheric coefficients A,B,C,D,E,F,G,H and the X-radius of curvature (except conic constant K) of surface 3 are picked up from surface 1. This is a group pickup, i.e. all aspheric coefficients (including CUX) are picked up from the designated surface (surface 1).
PIK D s	3 s1	Pick up aspheric coefficient $D$ only. Disables group pickup on s3, if previously enabled.
PIK GLA	s4 s1	As above, material properties of surface 5 are picked up from surface 1

### 8.15.1 Group Pickups

Individual pickups may be grouped together as a single entity. This holds for tilt/decenter pickups and asphere pickups only. Group pickups are entered in the command line by

PIK	DEC	s3	s1	Pickup all decenter/tilt parameter at surface 3 from surface 1 (group pickup)
PIK	ASP	s4	s2	Pickup all aspheric coefficients at surface 3 from surface 1 (group pickup)

In the surface editor, group tilt/decenter pickups are specified by selecting the "Decenter, Tilts" tab and entering the pickup surface in the "Pik" column, as shown in Fig. 8.22.

Individual pickups																
📢 Surface Editor: E:\optalix\examples\Misc\DOUBLE_GAUSS.OTX																
Standard Data	Decenter, Tilt:	S Asphe	re GRIN	Solve	es   Special Apert	ures	-	Hologram   Mis	SC.	1						
	THR	TLM	SEQ.	Pik	XDE			YDE		ZDE		ADE		BDE		
OBJS	0.00000	DAR	XYZABC		0.00000	Π		0.000000		0.00000	)	0.00000	Π	0.000000	Т	-
1 S	0.00000	DAR	XYZABC		0.000000		7	0.000000		0.00000	)	0.00000		0.000000	T	
2 AD	0.00000	DAR	XYZABC		3.000000		ļ	4.000000		0.000000		0.00000		0.000000	T	-
3 SDA	0.00000	DAR	XYZABC	2	6.000000	2		8.000000	2	0.00000	) 2	0.00000	2	0.000000	2	
STO AD	0.00000	DAR	XYZABC	1	0.000000			3.000000	П	0.000000		0.00000		0.000000	T	-
IMG S	0.00000	NAX	XYZABC		0.000000			0.000000	Π	0.00000	)	0.00000		0.000000		
									_						Þ	

Group pickup

Figure 8.22: Defining group pickups for tilt/decenter parameter.

Note that individual pickups (shown in the columns right to each parameter column) reflect the setting of the group pickup. Specifying an individual pickup (see sect. 8.15.3) will automatically remove the group pickup on that particular surface.

# 8.15.2 Individual Pickups

Individual pickups are applicable only for tilt/decenter parameters and aspheric parameters. An individual pickup specifies a pickup for a single parameter only. For example,

PIK E s3 s1	Pickup only E aspheric coefficient at surface 3 from surface
	1 (individual pickup)
PIK YDE s3 s1	Pickup only YDE decenter value at surface 3 from surface
	1 (individual pickup)

Entering an individual pickup will automatically remove the group pickup on that particular surface.

Individual pickups																
Standard Data	Decenter, Tilt	S Aspher	e GRIN	Solv	es Special Apert	ure	s	Hologram	lisc.					,	-	
	THR	TLM	SEQ.	Pik	XDE			YDE		<b>X</b> DE		ADE		BDE		<u></u>
OBJ S	0.00000	DAR	XYZABC		0.000000		7	0.00000	λ.	0.000000	Т	0.000000	Т	0.000000	Т	-
1 S	0.00000	DAR	XYZABC		0.00000		/	0.00000	)d	1.000000		0.000000		0.000000		_
2 AD	0.00000	DAR	XYZABC		3.000000	7		4.00000	)0	0.00000		0.000000		0.000000		_
3 SDA	0.00000	DAR	XYZABC		3.000000	2		-4.00000	)0 ·2	1.000000	1	0.000000		0.000000		_
STO AD	0.00000	DAR	XYZABC		0.00000			3.00000	)0	0.000000		0.000000		0.000000		_
IMG S	0.00000	NAX	XYZABC		0.000000			0.00000	)0	0.000000		0.000000		0.000000		
					$\mathbf{h}$											Þ

Group pickup not specified (enter 0 or blank)

Figure 8.23: Defining individual pickups for tilt/decenter parameters.

## 8.15.3 Pickups vs. Solves

Pickups are evaluated prior to solves. That is, a solve on the same surface affecting the pickup parameter will override the pickup value. Consider the following example:

cpi s3 1 sol umy s3 -0.1

The first command cpi s3 1 picks the curvature on surface 3 from surface 1. The second command, however, alters (solves) the curvature on surface 3 such that the paraxial marginal ray angle on surface 3 is -0.1. The pickup on surface 3 will be ineffective.

Note that aperture data cannot be picked up. This is due to multiple apertures being allowed on a surface.

## 8.15.4 Listing Pickups

Listing pickups is accomplished by the command LIS PIK. Here is a sample output:

PICK	UPS :				
#				Factor	Offset
2	PIK	DEC	3	1.0000	0.0000
3	PIK	CUY	2	0.0000	0.0000
3	PIK	ASP	2		
3	PIK	THI	1	0.0000	0.0000
3	PIK	GLA	1		
# 8.16 Solves

In contrast to linked (pick-up) surfaces, which only affect surface parameters, solves allow control of paraxial properties. Conditions for specifying a solve are, for example, holding the paraxial ray angle, the paraxial ray height or a certain paraxial ray incidence angle to a specified value. Solves will keep these requirements satisfied. For example, a paraxial ray angle solve at a surface will change its radius of curvature to maintain the specified ray angle. It is to be noted, that solves only apply to *paraxial* quantities. In optimization, this also makes it possible to reduce the number of independent variables.

	Sets a solve at surface sk. solve_type can be any 3-character		
	string of		
	UMX	solve x-curvature on sk to produce a ray exit angle	
	UMY	solve y-curvature on sk to produce a ray exit angle	
	HMX	solve axial separation/thickness on sk to produce a paraxial height param1 in the X/Z-plane at surface sk+1.	
	HMY	solve axial separation/thickness on sk to produce a paraxial height param1 in the Y/Z-plane at surface sk+1.	
SOL sk solve_type param1 param2	UCY	Solve paraxial direction angle (in radians) of the chief ray at surface(s) sij and zoom position zij with reference to a nominal input field angle of 1.0	
	НСҮ	Solve paraxial height of the chief ray at surface(s) sij and zoom position zij	
	AMY	solve Y-curvature on sk to make it aplanatic to the paraxial marginal ray.	
	IMY	solve Y-curvature on sk for an angle of incidence (param1) of the marginal ray. (param2) is not used.	
	ET	solve axial thickness on sk for an edge thickness (param1) at semi-diameter param2.	
	Delete so	lve of solve_type at surface sk.	
DEL SOL sk solve type	Example	:	
Dill Soll Sk Solveltype	DEL SO	l S4 UMY	
LIS SOL [sij]	List solves		
PIM yes no			
	Paraxial image solve. yes adjusts the back focal distance to the <i>paraxial</i> image location, no keeps the back focus fixed.		
		continued on next page	

continued from previous page	
RED reduction_ratio	Reduction ratio solve. Dynamically (i.e. as the optical system changes) set the paraxial object distance required to satisfy
	$RED = \frac{ImageHeight}{-ObjectHeight} = -m \tag{8.48}$
	where $m$ is the optical magnification. For an object at infinity $m = 0$ , any other value establishes a finite conjugate system. See also the SET MAG command on page 44, which adjusts magnification statically (i.e. one-time adjustment) and the notes below.
DEL RED	Delete solve on reduction ratio. Leaves object distances un- solved.

### **Examples:**

sol	umy s3 -0.1	Solve curvature at surface 3 to produce a marginal ray angle of -0.1 (radians).
sol	s3 et 0.1 15	Solve axial thickness at s3 such that an edge thickness of 0.1mm is achieved at a radial surface height of 15 mm.
sol	et s4 0 15	Solve axial thickness at surface 4 for 0mm edge contact at a semi- diameter 15mm.
red	2.0	Solves for object distance to satisfy optical magnification -2.0.
pim	У	Solves for paraxial image.

#### Notes:

- In zoomed systems, solves only apply to the first zoom position. The resulting value is then used in all zoom positions.
- In finite conjugate systems, the system aperture should be defined by the entrance pupil diameter (EPD) or the stop surface semi diameter only. Avoid system aperture definitions like FNO or NA.
- In finite conjugate systems, the system aperture should be defined by the numerical aperture object (NAO) or the stop surface semi diameter only.
- A paraxial height solve (HMY) at the last surface (in order to hold the back focus) must not be used in conjunction with PIM, as PIM always sets the image surface to the paraxial focus, thus overriding the HMY solve.
- A paraxial height solve (HMY) should not be used in conjunction with a distance pick-up DPI. The height solve will always override the corresponding distance pick-up.
- A paraxial angle solve (UMY) should not be used in conjunction with a curvature pick-up CPI. The angle solve will always override the corresponding curvature pick-up.
- In optimization, solve parameter must not be used as a constraint. For example, a UMY solve and a UMY constraint at the same surface will add to the computing load and the constraint will be ignored.

• A RED solve is not accepted if paraxial ray solves are simultaneously set in the system. Exception: ET solve (edge thickness).

Solves will be updated each time a paraxial ray trace is required. The selected parameters (curvature, separation, ...) are forced to be dependent variables on system parameters, which are solved directly. No iteration is required. Referring to the paraxial quantities in Fig.5.5, the relevant equations are for paraxial marginal ray angle (UMY = u'), solving for curvature c,

$$c = -\frac{u' - u}{(n' - n)h_a}$$
(8.49)

for paraxial marginal ray height at the subsequent surface (HMY = h'), solving for axial separation d,

$$d = \frac{h' - h}{u} \tag{8.50}$$

for a planatic condition (AMY), solving for curvature c

$$c = \frac{\left(\frac{1+n'}{n}\right) \cdot u}{h} \tag{8.51}$$

for angle of incidence (IMY = i), solving for curvature c

$$c = -\frac{i+u}{n \cdot h} \tag{8.52}$$

## 8.17 Tilted and Decentered Surfaces

The default condition is a centered system in which all surfaces are aligned along the optical axis. However, optical surfaces can be positioned arbitrarily in 3-D space. This is accomplished by tilting and/or decentering the coordinate system, in which the surface is described. The position of this coordinate system is specified by the XDE, YDE and ZDE parameters, its orientation is specified by the ADE, BDE and CDE parameters. By default, the positions/orientations of the (local) surface coordinate systems are always defined with respect to the global coordinate system (see DAR surface, section 8.18.1). Other forms of defining the local coordinate systems of subsequent surfaces are NAX (new axis) and BEN (bend at mirror). Tilt values are understood in a mathematical sense, i.e. positive tilts are counter clockwise (see also section 5.2.3 for a detailed definition of tilt orientation).

Tilts and decenter are non-commutative operations, i.e. tilting, then decentering results in a different coordinate system from decentering and then tilting. It is therefore important to specify the order in which tilts and decenter are applied to surfaces. The default condition is decenter first and then tilt.

ADE [sij sk] [zij zk]	Tilt angle (in degree) around X-axis . Positive tilts are		
alpha_tilt	counter clockwise.		
BDE [sij] [zij zk]	Tilt angle (in degree) around Y-axis. Positive tilts are		
beta_tilt	counter clockwise.		
CDE [sij] [zij zk]	Tilt angle (in degree) around Z-axis. Positive tilts are		
gamma_tilt	counter clockwise.		
XDE [sij] [zij zk]	X-decenter		
x_dec			
continued on next page			

continued from previous page	
YDE [sij] [zij zk]	Y-decenter
y_dec	
ZDE [sij] [zij zk]	
z_dec	Z-decenter
GADE [sij]	GRIN tilt around X-axis (This is an "ADE"-tilt of the GRIN
	material axis with respect to the surface vertex).
GBDE [sij]	GRIN tilt around Y-axis (This is a "BDE"-tilt of the GRIN
	material axis with respect to the surface vertex).
GCDE [sij]	GRIN tilt around Z-axis (This is a "CDE"-tilt of the GRIN
	material axis with respect to the surface vertex).
TLT sij	Tilt surface range sij. This command tilts a group of
	surfaces. The tilt angles and reference points are requested
	in a dialog box.
	Tilt mode, describes how the optical axis is defined after
	<pre>surface(s) sij:</pre>
	mode = $0$ : local decenter, (decenter and return, see DAR
	below.)
	mode = 1 : surface normal defines new optical axis, see
	NAX
TLM [sij]	mode = 2 : optical axis follows law of reflection at mirror
mode   DAR   NAX   BEN	(see BEN)
	Alternativaly, the tilt made may be entered by the same
	sponding acconving. For example
	TIM of NAX
	TIM 64 DEN atc
	Tilt sequence (order in which the decenter/tilt operations
	are applied) sequence is a character string of up to 6
	characters. The permitted characters are:
	X = decenter-X
	Y = decenter - Y
	Z = decenter-Z
TSEO [si i] soguence	A = tilt about X-axis
ISEQ [SI]] Sequence	B = tilt about Y-axis
	C = tilt about Z-axis
	The converse of tilt/dependence executions is enabled by the
	The sequence of the characters. For example, BV merful
	sequence of the characters. For example, BA performs the
	about 1-axis first, then decenter in A-direction. A YZABC
	is the default setting (i.e. decenter first, then tilts).
	continued on next page

continued from previous page	
TMAT sij sk glb_ref param112	Define surface decenter and tilt by a transformation ma- trix $M_{i,j}$ . The coordinate transformation may be referred to the coordinate system of a previous surface defined by glb_ref. Enter 0 for reference to the immediately pre- ceding surface. Twelve parameters param112 define the elements of the transformation matrix $M_{i,j}$ . The matrix elements $m_{i,j}$ are entered row wise. An example is given in sect. 8.20.1. For a detailed description of transforma- tion matrices see also section 8.20, page 116. Hint: Global transformation matrices defined in the system may be listed by the GSM command (page 183).
DAR [sij]	Surface decenter and return (equivalent command is TLM 0).
BEN [sij]	Surface bend, the optical axis follows the law of reflection at mirror (equivalent command is TLM 2).
NAX [sij]	New optical axis. The surface normal defines the new opti- cal axis for all subsequent surfaces (equivalent command is TLM 1).

## Notes:

Surface decenter and/or tilts only take effect if a surface type qualifier "D" is specified to the surface type. For example, a spherical tilted/decentered surface is set by the command SUT s3 SD. See also section 8.6 on page 68 for further details on surface types.

Consequently, tilts and/or decenter are deactivated for a particular surface by removing the "D" qualifier from the surface type string.

Unlike CODE V, DAR is the default tilt mode in OpTaliX.

Paraxial analysis may not be correct for non-symmetric systems, since the paraxial ray trace (by definition) does not account for decenters and tilts.

## 8.17.1 Sign convention for tilted surfaces:

The tilt angles ADE, BDE, CDE are referred to rotations around the X-, Y- and Z-axis respectively. The sign of the tilts follows the mathematical convention, i.e. a positive sign means a counter-clockwise rotation, a negative sign is a clockwise rotation (see Fig. 5.1 on page 30).

# 8.18 Tilt Modes

The method of tilting and decentering surfaces is specified by the tilt mode. Three types of decentered and tilted surfaces are provided. They can be specified by the following commands:

	Define the tilt-mode of surface (surface range) sij, where	
TIM si i tilt mode	<pre>tilt_mode = 0 : The optical axis is not changed (see also DAR command), tilt_mode = 1 : The new optical axis is the surface normal</pre>	
	of the actual surface (see NAX command),	
	tilt_mode = 2 The new optical axis follows the light path on	
	reflection on a mirror surface, without requiring an additional	
	tilted dummy surface. (see BEN command). To be used only	
	for mirror surfaces !!	
BEN sij	Bended surfaces. The new axis follows the law of reflection.	
	See detailed description in section 8.18.3	
DAR sij	Decenter and Return. See detailed description in section 8.18.1	
NAX sij	New axis. See detailed description in section 8.18.2	

The following sections give a more detailed explanation on the definition of tilt modes.

## 8.18.1 Tilt Modus 0 : Decenter and Return (DAR)

The "decenter and return" surface (Tilt modus = 0) is the default for tilted and decentered surfaces in OpTaliX. This option means that if a decentered surface is specified (either by DAR or TLM command), the subsequent surfaces refer to the coordinate system of the surface of the last TLM = 1 or TLM = 2 specifier. Example (Fig. 8.24):



Figure 8.24: Definition of tilted/decentered surface with tilt mode (TLM) = 0

Surface 3 is decentered and tilted by the following command sequence:

SUT	S3	SD	! surface type is spheric and decentered
TLM	s3	0	! Tilt modus is 0 (not initially required because TLM 0 is the default,
			however, if the surface is in a different tilt mode (1 or 2), then this com-
			mand must be explicitly given to set the surface to this mode).
DAR	s3		Decenter and return surface. This command is synonymous to "TLM
			s 3 0" as given above.
YDE	s3	2.5	! Y-decenter of surface 3 is +2.5mm
ADE	s3	30.	! Tilt around X-axis is 30 deg (counter clockwise since tilt is positive).

The subsequent surface 4 lies on the optical axis again, since surface 3 does not alter the optical axis. If a previous surface (for example surface 2) is a surface with TLM=1 or TLM=2, surface 4 (in the example of Fig. 8.24) refers to the previous surface surface 2). DAR-surfaces ("decenter and return")

need not to be initially specified (since they are the default) but they may be explicitly forced by :

TLM si..j 0 or DAR si..j

#### 8.18.2 Tilt Modus 1 : Surface Normal defines new Axis (NAX)

The tilt modus 1 (see TLM command) applied to a surface  $s_x$  sets the coordinate system for all subsequent surfaces to the local coordinate system of the surface  $s_x$ . The new optical axis coincides with the normal of surface  $s_x$ . The command sequence to generate the configuration of Fig. 8.25 is:

SUT S3 SD! surface type is spheric and decenteredTLM s3 1! Tilt modus is 1 (axis follows normal of preceding surface)YDE s3 2.5! Y-decenter of surface 3 is +2.5mmADE s3 30.! Tilt around X-axis is 30 deg (counter clockwise since tilt is positive).



Figure 8.25: Definition of tilted/decentered surface with tilt mode (TLM) = 1, i.e. the optical axis follows surface normal of the preceding surface.

#### 8.18.3 Tilt Modus 2 : Bend Surface (BEN)

The optical axis follows the reflection by a mirror. The ADE, BDE tilts are applied a second time after reflection in order to generate the new optical axis (see Fig. 8.26).

#### 8.18.4 Compound Tilts on a BENd Surface

A CDE tilt is automatically applied to compound tilts (ADE and BDE) on BEN type surfaces to keep the coordinate system properly applied. This rotates the system following a BEN surface so that a meridional ray will remain a meridional ray in the surfaces following the BEN surface. OpTaliX generates the CDE, it cannot be entered manually. The relationship between CDE and (ADE, BDE) is

$$\cos(CDE) = \frac{\cos(ADE) + \cos(BDE)}{1 + \cos(ADE)\cos(BDE)}$$
(8.53)



Figure 8.26: Definition of tilted/decentered surface with tilt mode (TLM) = 2, i.e. optical axis follows law of reflection.

The calculated CDE is reported in the prescription data (see LIS command). If CDE is explicitly required on a BEN surface (for example in non-rotationally symmetric systems), BEN should be removed from this surface and the corresponding decenters/rotations should be applied to an extra dummy surface.

## 8.18.5 Reverse Decenter and Tilts (REV)

The REV command takes the decenter/tilt information on a surface and applies the inverse.

REV [sij]	Takes decenter and tilts and applies it with inverse sign
	and reverse order.

# 8.19 Tilt Sequence

Any sequence of tilts and decenter may be specified. The default sequence is given in table 8.22.

Order	Tilt/decenter	Qualifier	Symbol
first	XDE (decenter X)	X	$\Delta x$
second	YDE (decenter Y)	Y	$\Delta y$
third	ZDE (decenter Z)	Z	$\Delta z$
fourth	ADE (tilt about X-axis)	A	$\alpha$
fifth	BDE (tilt about Y-axis)	В	$\beta$
sixth	CDE (tilt about Z-axis)	С	$\gamma$

Table 8.22: Default tilt sequence and qualifying characters.

The tilt sequence is specified by a 6-character string, describing the sequence of decenter/tilts. For the default sequence, the tilt sequence would be "XYZABC", which corresponds to decenters  $\Delta x$ ,  $\Delta y$ ,  $\Delta z$  and the Euler tilt angles  $\alpha$ ,  $\beta$ ,  $\gamma$ . This means, that decenters are applied before tilts. The tilt/decenter sequence is entered by the command

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TSEQ [sij] string	Tilt sequence. Specify the sequence of tilts or decen-
	ters by a 6-character string. The default sequence is
	XYZABC.

Unlike in other optical design programs, an arbitrary sequence not only allows changing the order of tilts and decenter (e.g. decenter-after-tilt or tilt-after-decenter), it also permits arbitrary sequences within tilts or decenters (e.g. first around Z-axis, second around X-axis, third around Z-axis) and even mixed sequences of decenters and tilts.

It is important to note, that the order of tilts and decenters matters. The tilt sequence  $\alpha, \beta, \gamma$  does not provide the same result as the tilt sequence  $\beta, \alpha, \gamma$  or  $-\alpha, -\beta, -\gamma$  with the same tilt/rotation angles, or any other arbitrary combination.

Tilting is performed internally by successive matrix multiplications, applied in the specified sequence. For example, the default tilt sequence (i.e. first tilt around X-axis, second around Y-axis, third around Y-axis) results in the following matrix multiplication (from right to left)<sup>1</sup>

$$M_{z} \cdot M_{y} \cdot M_{x} = \begin{bmatrix} \cos \gamma & \sin \gamma & 0 & 0 \\ -\sin \gamma & \cos \gamma & 0 & 0 \\ 0 & 0 & 1 & 0 \\ 0 & 0 & 0 & 1 \end{bmatrix} \cdot \begin{bmatrix} \cos \beta & 0 & -\sin \beta & 0 \\ 0 & 1 & 0 & 0 \\ \sin \beta & 0 & \cos \beta & 0 \\ 0 & 0 & 0 & 1 \end{bmatrix} \cdot \begin{bmatrix} 1 & 0 & 0 & 0 \\ 0 & \cos \alpha & \sin \alpha & 0 \\ 0 & -\sin \alpha & \cos \alpha & 0 \\ 0 & 0 & 0 & 1 \end{bmatrix}_{rotation \ around \ X}$$
(8.54)

In case of uncertainties, it is always possible to spread the tilts out over several dummy surfaces.

## 8.20 Transformation Matrix

Surface tilts and decenters may also be defined by so-called transformation matrices. A transformation matrix gives a unique representation of location and orientation of a surface with respect to another surface or to a global coordinate system. Surface matrices can be entered by the TMAT command. Before entering transformation matrices we shall be concerned with the definition of a transformation matrix which is a 3x4 matrix of the form

$$M_{i,j} = \begin{bmatrix} m_{1,1} & m_{1,2} & m_{1,3} & m_{1,4} \\ m_{2,1} & m_{2,2} & m_{2,3} & m_{2,4} \\ m_{3,1} & m_{3,2} & m_{3,3} & m_{3,4} \end{bmatrix}$$
(8.55)

A transformation matrix describes tilts and decenters of the vertex normals (i.e. the local coordinate system) of a surface with respect to another coordinate system which can be the coordinate system of a previous surface or of a global coordinate system.

Coordinate transformations are performed by tilts about the local X-axis ( $\alpha$ ), Y-axis ( $\beta$ ), Z-axis ( $\gamma$ ) and decenters (X, Y, Z). See also the definition of (local or global) coordinate systems in section 5.2, page 29. We also note that tilts are not commutative, that is, the order of tilts matters.

Tilt of a surface about the X-axis:

$$M_{i,j} = \begin{bmatrix} 1 & 0 & 0 & 0\\ 0 & \cos \alpha & \sin \alpha & 0\\ 0 & -\sin \alpha & \cos \alpha & 0 \end{bmatrix}$$
(8.56)

<sup>&</sup>lt;sup>1</sup>Only 3x4 matrices are needed to fully describe surface tilt and decenters. In OpTaliX these matrices are extended to 4x4 matrices. This is a marginal overhead but greatly simplifies matrix operations in a form suited for computers.

Tilt of a surface about the Y-axis:

$$M_{i,j} = \begin{bmatrix} \cos \beta & 0 & -\sin \beta & 0 \\ 0 & 1 & 0 & 0 \\ \sin \beta & 0 & \cos \beta & 0 \end{bmatrix}$$
(8.57)

Tilt of a surface about the Z-axis:

$$M_{i,j} = \begin{bmatrix} \cos\gamma & \sin\gamma & 0 & 0\\ -\sin\gamma & \cos\gamma & 0 & 0\\ 0 & 0 & 1 & 0 \end{bmatrix}$$
(8.58)

Lateral shift (decenter):

$$M_{i,j} = \begin{bmatrix} 1 & 0 & 0 & -X \\ 0 & 1 & 0 & -Y \\ 0 & 0 & 1 & -Z \end{bmatrix}$$
(8.59)

### Example:

A 20° tilt about the X-axis plus a 5mm decenter in Y-direction results in the transformation matrix

$$M_{i,j} = \begin{bmatrix} 1 & 0 & 0 & 0\\ 0 & 0.8660254 & 0.5 & -5\\ 0 & 0.5 & 0.8660254 & 0 \end{bmatrix}$$
(8.60)

## 8.20.1 Entering Transformation Matrices:

A 20° tilt about the X-axis plus a 5mm decenter in Y-direction is entered as follows:

tmat s4 0 1 0 0 0 0.8660254 0.5 -5 0 -0.5 0.8660254 0

This is a very cryptic form of entering a transformation matrix. So, it is advisable putting this command in a macro file which allows arrangement of the data in a matrix-like fashion for better readability. We define the following text in a file, say tmat.mac

tmat	s4	0	1.0000000	0.000000	0.000000	0.000000	&
			0.000000	0.8660254	0.5000000	-5.000000	&
			0.000000	-0.5000000	0.8660254	0.000000	

and execute the macro from the command line with

run tmat.mac

Note the operator for line continuation (&) in the macro example above. Hint: Global transformation matrices defined in the system may also be listed/controlled by the GSM command (page 183).

# 8.21 Tilting GRIN Material Properties

The alignment of the refractive index profile of GRIN materials is defined by the tilt mode of the surface, which specifies the GRIN material properties. By default, the GRIN profile is aligned along the optical axis, but it may be laterally and axially displaced using the GXDE, GYDE, GZDE commands or may be differently oriented using GADE, GBDE, GCDE commands. In addition, the tilt mode (DAR

or NAX) of the surface holding the GRIN material properties also affects the orientation of GRIN media. The combination of *surface* tilts/decenters and *GRIN* tilts/decenters can be a complicated process. Figs. 8.27 and 8.28 illustrate the absolute orientation of GRIN profiles for various tilt modes.



Figure 8.27: Orientation of GRIN profiles with DAR surfaces. Left: Since a DAR surface does not alter the optical axis, the index of refraction profile of the GRIN medium is also aligned along the optical axis. Right: Use GADE, GBDE, GCDE to tilt the GRIN profile with respect to the optical axis.



Figure 8.28: Orientation of GRIN profiles with NAX surfaces. Left: The vertex normal of a NAX surface defines the new optical axis. Thus, the profile of the GRIN medium is also aligned along the *new* optical axis. Right: Use GADE, GBDE, GCDE to additionally tilt the GRIN profile with respect to the *new* optical axis.

Note that BEN (bend) surfaces are not allowed in conjunction with GRIN media. If the bend function is explicitly required inside GRIN media, it should be applied to an extra dummy surface.

## 8.22 Global Referencing

Any surface may be referenced to the local coordinate system of a *previous* surface. In this manner it is possible to break the strict sequential order of surfaces (where the local coordinate system of a surface refers to its preceding surface), even though the ray trace is still sequential.

Referenced surfaces must always be NAX-surfaces, which means that a subsequent surface is referred to the local coordinate system of the referenced surface. On entering a surface reference, the tilt mode is automatically set to 1 (see NAX, TLM).

GLB Sij k	Global surface reference. Coordinate data (XDE, YDE, ZDE, ADE,					
	BDE, CDE) are interpreted for surface(s) i j with respect to the co-					
	ordinate system of a <i>preceding</i> surface k. Tilts and decentrations are					
	recalculated to retain the physical position of the surface. A surface					
	which is already globally referenced may be referenced to another					
	surface by simply reapplying the GLB command with the new (pre-					
	ceding) surface number. Global referencing can be removed by GLB					
	sij 0					
REF Sij k	Specifies a global reference for surfaces i j with respect to					
	surface k. The difference to the GLB command is that thick-					
	ness/tilt/decentration data are not altered. This may result in a change					
	of the optical layout. Warning: The "REF sij" command must					
	not be confused with the command "REF ref_w" which changes the					
	reference wavelength. Distinction is made by the surface qualifier					
	sij wether REF means a reference to another surface or the ref-					
	erence wavelength.					
THR sik ref_thi	$\mathbf{P} = \{\mathbf{r}_1, \dots, \mathbf{r}_k\}  \text{if } \mathbf{r}_1 = \mathbf{r}_1 + \mathbf{r}_2 + \mathbf{r}_1 + \mathbf{r}_2 + \mathbf{r}_1 + \mathbf{r}_2 + \mathbf{r}_2 + \mathbf{r}_1 + \mathbf{r}_2 + \mathbf$					
	Reference thickness of surface(s) 1 j to surface k is refithi. The					
	reference thickness is measured from the referenced surface (k) to the					
	referencing surface $(ij)$ . The referenced surface k must have a					
	lower number than the referencing surface i.					

To explain the concept of global referencing, let us consider a simple system with a moveable lens (see Fig. 8.29). Here, the image surface (surface 7) is referred to the local coordinate system of surface 1 instead of being referenced to its previous surface (surface 6), as would be expected in a strict sequential model. In this example, surface 7 is the *referencing* surface, surface 1 is the *referenced* surface. This is accomplished by two commands:

GLB	s7	1	! Surface 7 is referenced to surface 1
THR	s7	194.7	! The reference thickness of surface 7 to surface 1 is 194.7mm, i.e.
			surface 7 is 194.7mm separated from the local vertex of surface 1

Thickness 6 can no longer be freely altered by the user because it has become a *dependent* variable. Its value is computed from the thicknesses 1 to 5 and from the absolute position of surface 7 (the referencing surface). In the surface spreadsheet editor, the field for thickness 6 is greyed out. We note.

- The position of a globally referenced surface is solely determined by the THR value on this surface,
- THR is an *independent* variable and is always specified as the separation *before* the referencing surface,
- the thickness before a globally referenced surface is always a *dependent* variable (greyed out in the surface editor).

We also note that specifying the reference thickness THR as the separation *before* the referencing surface is in contrast to the convention used in OpTaliX (separations are always defined as distance from the local surface to the subsequent surface. Using this method, it is straightforward to change the separation between the doublet and the negative lens (thickness 4) without affecting the position of the image surface (as it would be in a model of strictly consecutive surface separations). Thus, we now have an elegant way to keep the overall length of the system constant without compromising or



Figure 8.29: Definition of surface references.

altering other system parameters. Such a feature is particularly useful in zoomed (multi-configuration) systems where only one parameter needs to be controlled, instead of two (the separation before and after a lens group). We will now move the negative lens by changing thickness 4: The position of the lens relative to surface 4 has changed while the image plane position remains the same, because it is referred to the vertex of surface 1 which has not changed (Fig. 8.30).



Figure 8.30: Definition of surface references.

From these considerations it is now evident, that a *referencing* surface has two axial thicknesses, THR and THI. While THR refers the vertex of a surface to the vertex of another (*previous*) surface, THI defines the thickness to the subsequent surface.

# 8.23 "No-Raytrace" (NOR) Surface

A "no-raytrace" (NOR) surface is a special surface that only transforms surface and ray coordinates, but does not actually trace rays to this surface. NOR surfaces are particularly useful for optical systems that contain tilts and decenters, however, they may also be favourably used in centered systems. NOR surfaces can be used to define non-optical reference points such as mechanical interfaces (flanges, polygon scanner rotation axis, etc) and refer optical surfaces and components to these points.

NOR surfaces require the surface type (SUT) "X", which is obligatory. The surface type qualifiers "S", "A" or "L" must not be contained in the surface type definition. The command

NOR si..j

does all the necessary actions to convert a surface to a "no-raytrace" (NOR) surface. NOR surfaces can be centered or decentered. Thus, NOR surfaces are only defined by the surface types "X" or "XD". Other surface types (such as the optional qualifiers M,I,H,G, ...) are allowed but have no effect on the ray trace.

Note that NOR surfaces do not return ray intersection data – for example as displayed in ray intersection plots (SPO RIS), single ray trace analysis (RSI) or in footprint analysis (FOO), because rays are not actually traced to the designated surface (only coordinates are transformed). Therefore, ray intersection coordinates cannot be made available on NOR-surfaces!

NOR surfaces, together with globally referenced surfaces, provide a powerful means for modelling opto-mechanical effects. Their use is explained on the example of a polygon scanner as shown in Fig. 8.31. We will use both global referencing and NOR surfaces to achieve the desired effect of moving polygon facets. In this model, surface 1 (the first surface of the  $F\theta$  - lens) is globally referenced to surface 1, the stop surface. Since the  $F\theta$  lens is tilted by 90° with respect to the entrance beam at surface 1, the desired position is accomplished by the commands

glo	s5	1	! global reference of surface 5 to surface 1. Surface 5 is automat-
			ically converted to decentered type with tilt mode NAX.
ade	s5	90	! tilt surface 5 by 90°
yde	s5	50	! Y-vertex position of surface 5
thr	s5	25	! reference thickness is 25mm, that is the Z-separation of the
			vertex of surface 5 from surface 1.

Surface 2 is located at the polygon's rotation axis. The Z-position (along the optical axis) is defined by THI s1, the Y-position is entered by a YDE s2 command. Surface 2 is of decenter type NAX, thus surfaces 3 and 4 refer to surface 2. Surface 3 is not really needed, it is only used in this example to better visualize the polygon center by plotting a cross. Surface 4 represents one mirror facet of the polygon. Its tilt and decenter values are appropriately set with reference to surface 2.

Note that the global decenter type on surface 5 avoids the need to apply a second tilt angle on a dummy surface to keep the geometry fixed.

Surfaces 2 and 3 are made NOR surfaces by the command NOR s2..3, thus avoiding that rays are apparently plotted "through" the polygon facet mirror (surface 4) to surfaces 2,3. Surfaces 2 and 3 are solely used for transformational purposes and need not to be traced by real rays.

# 8.24 Gradient Index Surface

In inhomogeneous or *gradient-index* materials, rays no longer propagate in straight lines. The index of refraction changes as a function of the position of the ray in the medium. A gradient in the direction of the optical axis is called an axial gradient, a gradient perpendicular to the optical axis is called a radial gradient. Of course, there are mixed gradients possible, in which the index of refraction is a function of axial and radial position in the material.

A complete specification of a gradient surface must take into account the surface properties as well as the material properties. The qualifier "I" must be added to the surface type to tell the program how refraction into the gradient-index material shall be performed. The material properties may be defined by either specifying a predefined gradient-index glass (e.g. G14SFN for Gradium<sup>TM</sup> glass) or by entering gradient coefficients for each of the defined wavelengths.

The numerical solution of finding the exact ray path involves the choice of a step size ds. Choosing small values for ds will improve numerical accuracy, however, will also increase computing time.



Figure 8.31: Use of global coordinates and NOR surfaces for modelling of a polygon scanner.

SUT sij string	Surface Type (SUT) of surface(s) i.j is "string". Note that		
	the surface type must contain at least a S (for spherical sur-		
	faces) or A (for aspheric surfaces) within string. Example: sut		
	s3 ai (aspheric + GRIN)		
	Glass name. The specification of the glass name takes prece-		
	dence over the base index specification . It automatically		
	causes proper setting of the base index and the gradient index		
	coefficients for all specified wavelengths. If glass name is		
	omitted, at least the base refractive index (i.e. refractive index		
	at the optical axis) must be given. There are predefined glasses		
GLA sij name	for the gradient types LPT, NSG and GLC (see GIT command		
	below). For all other types of gradients where the index profile		
	is defined by manual entry of coefficients (GIC), the generic		
	glass "GRIN" must be used. Examples:		
	gla s2 g41sfn (LightPath Gradium $^{TM}$ -glass)		
	gla s2 grin (generic GRIN-glass, enter coefficients		
	with GIC command)		
	continued on next page		

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continued from previous page	
GIC sij cij val	Gradient index profile coefficients. The definition of the coefficients c1, c2, c3, in dependence on the GRIN-type (GIT) is given in table 8.24.16. In order to take effect, the glass type (GLA) must be GRIN. Other gradient index glasses (for example G51SFN from LightPath or SLW18 from Nippon Sheet Glass Corp., etc.) have predefined profile coefficients, which cannot be changed.
GDISP sk disp_name	Gradient index dispersion name. Defines which user defined dispersion characteristics is assigned to a gradient index ma- terial on surface sk. Note that the glass type (see GLA com- mand) on surface sk must be GRIN. This command does not work with predefined gradient index materials. The disper- sion coefficients are defined in the file grindisp.asc in the GLASSES directory and are then globally available. See also section 32.9 for a definition of the file format. Currently only LPT, URN, SEL, GLC and GRT dispersion models may be se- lected. If disp_name is left blank, dispersion properties are removed from the GRIN material on surface sk.
GIS sij step	Gradient step size $ds$ . The parameter step is the integration step along the ray path. See also the note at the end of this table.
GZO sij val	Gradient Z-offset, for axial gradients only. Describes the axial offset of the vertex of the entrance surface from the zero-point of the axial index function.
GADE [sij] val	GRIN tilt around X-axis (This is an "ADE"-tilt of the GRIN material axis with respect to the preceding surface).
GBDE [sij] val	GRIN tilt around Y-axis (This is a "BDE"-tilt of the GRIN ma- terial axis with respect to the preceding surface).
GCDE [sij] val	GRIN tilt around Z-axis (This is a "CDE"-tilt of the GRIN ma- terial axis with respect to the preceding surface).
GIT sij string	Gradient Index Type. The following types of gradient index profiles are available:         SEL :       SELFOC gradient         GLC :       Gradient Lens Corporation Gradient (EndoGRIN <sup>TM</sup> )         GRT :       Radial gradient from Grintech, Jena         LPT :       LightPath GRADIUM axial gradient         AXG :       Linear axial gradient         URN :       University of Rochester gradient         LUN :       Luneberg Lens         SPG :       Spherical gradient         MAX :       Maxwell's Fisheye         Example: git s3 lpt ! LightPath Gradium <sup>TM</sup> -glass
	continued on next page

continued from previous page	
MXG sij sk max_grin_iterations	Maximum number of iteration steps in the GRIN medium de- fined on surface(s) sij sk. Gradient index ray trace may loop infinitely if improper coefficients are specified, in particu- lar for user defined profiles. Note that each gradient index sur- face may be assigned a different value for MXG. Setting MXG to values other than 0 provides a means to prematurely termi- nate ray tracing. MXG sij sk 0 disables limit checking on that particular surface(s).

Note on optimal gradient-index step (GIS): The accuracy and speed of gradient-index ray tracing is determined by the choice of step length. The default step size in OpTaliX is set to 0.1 mm, which is a good compromise for various gradients. It is recommended to test the step size until an acceptable accuracy is achieved for a particular system and, if required, to be reduced accordingly. As a guideline, the step size may be as large as 1mm for weak gradients without the need to sacrifice accuracy in geometrical analysis. For diffraction analysis, however, typically smaller step sizes are required for acceptable accuracy. In cases, where a large step size (> 0.1mm) is selected, the program automatically reduces step size to 0.1mm in all diffraction analyses and restores the user selected step size afterwards.

Aperture checking for gradient index surfaces may be accomplished by assigning the fixed aperture flag FHY (see section 8.33.3) on the first surface of a GRIN lens. Rays inside the gradient material are blocked if their radial coordinate exceeds the aperture of the entrance surface.

#### **Example Commands:**

SUT	s3	AI	! surface type of surface 3 is AI (aspheric, gradient index)
GLA	s3	SLN20	! glass type at surface 3 is SLN20
GIT	s3	SEL	! gradient index type at surface 3 is SEL (=SELFOC lens)
GIC	s3	c4 0.42	! gradient index coefficient No.4 = $0.42$ for all wavelengths
GZO	s3	1.2	! gradient z-offset = 1.2 mm
MXG	s3	200	! Limit number of iterations in GRIN medium defined on surface
			3 to 200.

## Example 1: Setting up a LightPath GRADIUM $^{TM}$ gradient:

Defining LightPath GRADIUM<sup>TM</sup> gradients only requires specification of the LightPath glass name, e.g.

GLA s2 G14SFN

All other parameters (gradient index type, surface type) are automatically determined. In addition, when switching back from a LightPath GRADIUM glass to a homogeneous glass, the gradient index type and the surface type are automatically reset.

### **Example 2: Defining gradient material with coefficients:**

If a predefined gradient material does not exist or if a user profile shall be simulated, the index profile may be defined by entering profile coefficients directly. The coefficients depend on the gradient type chosen, as explained in Eq's. 8.67 to 8.86 and in table 8.24.16 (page 132).

For example, a "University of Rochester (URN)" gradient consists of axial and radial coefficients, thus allowing definition of a mixed gradient.



Figure 8.32: Gradient index raytrace, shown for a radial index profile.

gic	s3	c1	1.65	defines $1^{st}$ profile coefficient (the base index $n_{00}$ )
gic	s3	c2	-0.035	defines $2^{nd}$ profile coefficient (the linear axial slope $n_{01}$ )

## 8.24.1 Editing GRIN Coefficients on a Surface

In addition to selecting own GRIN dispersion models via the GDISP command, coefficients may also conveniently edited in a dialog called from the surface editor. The major difference to the GDISP option is that the GRIN material is only defined on a particular surface in a lens and is therefore not globally available as with predefined GRIN materials.

In order to enable this option, the glass name on the surface must be 'GRIN'. No other name is allowed. Then select the GRIN-tab in the surface editor and click on the appropriate button in the 'Coeff' column. This opens a dialog as shown in Fig. 8.33. You may now select a predefined dispersion characteristics (as defined in '\$ i\glasses\grin.asc' for catalogue GRIN's or in '\$ i\glasses\grin.asc' for catalogue GRIN's or in '\$ i\glasses\grin.asc' for user defined dispersions) or you may select the 'USER' option in the list box. If 'USER' is selected, the dispersion coefficients can be edited, otherwise (for predefined dispersions) the coefficients field is disabled (greyed out). The name 'USER' in the list box may be changed at wish.

'User' defined profiles and dispersions always pertain to the particular surface from which the dialog was called. The 'USER' definitions are stored with the optical system and are therefore only 'locally' available within that particular optical system.

	Profile Coefficient	Dis	persion Name	JSER		•
z_max	13.93126					10
n_0	1.738380	IVIII	i. wavei. j 0.3		waver j 0.130	
n_1	-0.2782390E-01	Rel	f. Wavel.   0.5	876		
n_2	0.2659603	Kr	max f			<u> </u>
n_3	-7.178033		I			<u> </u>
n_4	63.22996		i=1	i=2	i=3	
n_5	-307.9833	K1i	0.52266E-02	0.20698E-01	-0.45030E-02	
n_6	908.7213	K2i	0.47284E-01	0.42940E-01	-0.72488E-02	
n_7	-1686.475	K3i	0.98860	0.57962E-01	0.94167E-01	—
n_8	1980.927	L1i	0.42163E-01	0.0000	0.0000	—
n_9	-1429.700	L2i	0.36859E-01	0.0000	0.0000	—
n_10	578.8313	L3j	110.00	0.0000	0.0000	—
n_11	-100.6775					
	<b>~</b>					▶

Figure 8.33: Editing GRIN coefficients on a particular surface.

**Warning:** Altering GRIN coefficients should be done with great care. In case of improper data, the program may hang in an infinite loop because no exit surface is found. It is prudent to reduce the

maximum allowable number of GRIN steps on a surface before testing or experimenting with new profiles. See the MXG command.

#### 8.24.2 Ray-Tracing Method

Tracing rays in inhomogeneous (gradient) index material is obtained by solving the ray equation [49] :

$$\frac{d^2\mathbf{r}}{dt^2} = n\nabla n \tag{8.61}$$

with

$$t = \int \frac{ds}{n}; \qquad dt = \frac{ds}{n} \tag{8.62}$$

where  $\mathbf{r}$  is the position vector of a point on the ray, ds is an element of the arc along the ray. Equation 8.61 has three components which can be solved simultaneously by using three-element arrays:

$$\mathcal{R} \equiv \begin{pmatrix} x \\ y \\ z \end{pmatrix}$$
(8.63)

$$\mathcal{T} = \begin{pmatrix} T_x \\ T_y \\ T_z \end{pmatrix} = n \begin{pmatrix} dx/ds \\ dy/ds \\ dz/ds \end{pmatrix}$$
(8.64)

and

$$\mathcal{D} = n \begin{pmatrix} \frac{\partial n}{\partial x} \\ \frac{\partial n}{\partial y} \\ \frac{\partial n}{\partial z} \end{pmatrix}$$
(8.65)

It is obvious that the components of the vector  $\mathcal{T}$  are the three optical direction cosines  $\alpha, \beta, \gamma$  of a ray. Equation 8.61 can be written as the following matrix equation:

$$\frac{d^2 R}{dt^2} = \mathcal{D}(\mathcal{R}) \tag{8.66}$$

Equation 8.66 is solved by the Sharma method [49] with the initial condition that at  $\mathcal{R} = R_0(x_0, y_0, z_0)$ ,  $\mathcal{T} = T_0$  which is a known quantity. Starting from the known point  $(R_0, T_0)$ , one can generate successively  $(R_1, T_1), (R_2, T_2), \cdots , (R_n, T_n)$ , i.e., one can trace a ray through the medium using the *Runge-Kutta* algorithm.

### 8.24.3 SELFOC<sup>TM</sup> Lens (SEL)

The radial gradient of SELFOC<sup>TM</sup> lenses is given by:

$$n(r) = n_0 \left(1 - \frac{A}{2}r^a\right) \tag{8.67}$$

with

$$a = 2$$

$$A = \frac{2 \cdot \Delta n}{n_0 \cdot r_h^a}$$
(8.68)

In SELFOC<sup>TM</sup> material the refractive index decreases *parabolically*, which is defined by a = 2 in eq. 8.67. Substituting eq. 8.68 into eq. 8.67, we obtain, after some simple manipulations, the more general form

$$n(r) = n_0 - \underbrace{\frac{2 \cdot \Delta n}{n_0 \cdot r_k^a}}_{A} \cdot \frac{n_0 r^a}{2}$$
(8.69)

See also section 13.7.4 for a list of available GRIN profiles from NSG.

The wavelength dependency (dispersion) of SELFOC<sup>TM</sup> glasses is given by the equations [39]

$$n_0(\lambda) = c_1 + \frac{c_2}{\lambda^2}$$
 (8.70)

$$\sqrt{A}(\lambda) = k_{11} + \frac{k_{12}}{\lambda^2} + \frac{k_{13}}{\lambda^4}$$
(8.71)

#### 8.24.4 Gradient Lens Corporation (GLC)

The radial gradient of "EndoGRIN" rod lenses provided by "Gradient Lens Corporation" is:

$$n(r) = n_{00} + n_{10}r^2 + n_{20}r^4$$
(8.72)

where  $r^2 = x^2 + y^2$ .

The coefficients  $n_{00}$ ,  $n_{10}$ ,  $n_{20}$  are wavelength dependent:

$$n_{ij}(\lambda) = A + B\lambda^2 + \frac{C}{\lambda^2} + \frac{D}{\lambda^4}$$
(8.73)

where  $\lambda$  must be given in nm. For each  $n_{00}$ ,  $n_{10}$ ,  $n_{20}$  there exist a separate set of parameters A, B, C, D. See also section 13.7.4 for a list of available GRIN profiles from Gradient Lens Corp.

#### 8.24.5 Grintech Radial Gradient (GRT)

The radial gradient profile of rod lenses manufactured by Grintech, Jena (Germany) is defined as

$$n(r) = n_0 \cdot sech(gr) = \frac{n_0}{\cosh(gr)}$$
(8.74)

where  $r^2 = x^2 + y^2$  and g is a material constant. The dispersion of  $n_0$  is modelled with good accuracy by

$$n_0(\lambda) = 1.61189 + \frac{7614[nm^2]}{\lambda^2}$$
(8.75)

See also section 13.7.4 (page 234) for a list of available GRIN profiles from Grintech.

### 8.24.6 Grintech Cylindrical Gradient (GRC)

The gradient profile of cylindrical lenses manufactured by Grintech, Jena (Germany) is defined as

$$n(y) = n_0 \cdot sech(g \cdot y) = \frac{n_0}{\cosh(g \cdot y)}$$
(8.76)

where y is the height in Y-direction and g is a material constant. In the X-direction, the g-coefficient is assumed zero and the index of refraction is  $n_0$ . The dispersion of  $n_0$  is modelled with good accuracy by

$$n_0(\lambda) = 1.61189 + \frac{7614[nm^2]}{\lambda^2} \tag{8.77}$$

See also section 13.7.4 (page 234) for a list of available GRIN profiles from Grintech.

#### 8.24.7 Linear Axial Gradient (AXG)

The refractive index is a linear function of the axial distance z:

$$n(z) = n_0 + a \cdot z \tag{8.78}$$

with :  $n_0$  = base index at the optical axis a = linear axial coefficient

#### 8.24.8 LightPath Technologies Gradient (LPT)

LightPath Technologies, Inc. are using a  $11^{th}$  order axial profile for their proprietary GRADIUM<sup>TM</sup> glasses:

$$n(z) = \sum_{i=0}^{11} n_i \left(\frac{z}{z_m}\right) = n_0 + n_1 \left(\frac{z}{z_m}\right)^1 + n_2 \left(\frac{z}{z_m}\right)^2 + n_3 \left(\frac{z}{z_m}\right)^3 + n_4 \left(\frac{z}{z_m}\right)^4 + \dots + n_{11} \left(\frac{z}{z_m}\right)^{11}$$
(8.79)

where the coefficients  $n_0$  to  $n_{11}$  are given in ascending order at the wavelength  $\lambda_{ref} = 587.6nm$ . z is the distance into the blank from either the high index or low index surface. The value of z ranges from 0 to the maximum value  $z_m$ .

The wavelength dependence is modelled by a modified Sellmeier formula

$$n(\lambda)^2 - n(\lambda_{ref})^2 = \sum_i \frac{K_i \lambda^2}{\lambda^2 - L_i}$$
(8.80)

where  $n(\lambda_{ref})$  is the index at the reference wavelength and the constants are functions of n

$$K_{i} = \sum_{j=1}^{k} K_{ij} \left[ n(z, \lambda_{0}) \right]^{j-1}$$
(8.81)

and

$$L_{i} = \sum_{j=1}^{k} L_{ij} \left[ n(z, \lambda_{0}) \right]^{j-1}$$
(8.82)

The wavelength  $\lambda$  is given in microns. See also section 13.7.4 for a list of available GRIN profiles from LightPath Inc.

#### 8.24.9 University of Rochester Gradient (URN)

 $n(r,z) = n_{00} + n_{01}z + n_{02}z^2 + n_{03}z^3 + n_{04}z^4 + n_{10}r^2 + n_{20}r^4 + n_{30}r^6 + n_{40}r^8$ (8.83)

with :

 $r(x, y)^{2} = x^{2} + y^{2}$   $n_{00} = \text{base index}$   $n_{0i} = \text{axial coefficients}$   $n_{i0} = \text{radial coefficients}$ 

Dispersion properties can be assigned to URN gradient index profiles by specifying a *dispersion name* as provided in the GDISP command. The same set of dispersion coefficients as for the LightPath material is used. In particular Eqs. 8.80 to 8.82 apply. Dispersion coefficients must be stored in the file grindisp.asc in the GLASSES directory.

Example for setting up a generic URN profile with dispersion modelling:

gla	s1	GRIN	! generic name for gradient index glass
git	s1	URN	! gradient index type is URN
gic	s1	cl 1.678	! first profile coefficient
gic	s1	c2 0.00345	! second profile coefficient
gic			! repeat coefficients entry if required
gdis	sp s	s1 GLAK	! the dispersion name is GLAK (must exist in file grindisp.asc).

#### 8.24.10 Luneberg Gradient (LUN)

$$n^{2}(p) = n_{0}^{2} \left(2 - \frac{p^{2}}{a^{2}}\right)$$
(8.84)

with:  $p^2 = x^2 + y^2 + (z - r)^2$ 

### 8.24.11 Spherical Gradient (SPG)

$$n(p) = n_0 + n_1(r-p) + n_2(r-p)^2 + n_3(r-p)^3 + n_4(r-p)^4$$
(8.85)

with:  $p^2 = x^2 + y^2 + (z - r)^2$ 

#### 8.24.12 Maxwells's Fisheye (MAX)

$$n(p) = \frac{n_0}{1 + \frac{p^2}{a^2}}$$
(8.86)

with:  $p^2 = x^2 + y^2 + (z - r)^2$ 

1

## 8.24.13 User-Defined Gradient Index (UDG)

User-defined gradient index profiles can be programmed in FORTRAN or C in a user-written subroutine. The default name for a user-defined gradient index profile is "usergrn".

The usergrn subroutine must compute the refractive index at any point (x,y,z) in the glass, i.e., n = n(x, y, z). The subroutine must also explicitly evaluate the derivatives of the index, dn/dx, dn/dy, and dn/dz.

Coefficients of a user-defined gradient are specified by the UDG command:

UDG sij sk cij ck	
coeff_1 coeff_2	Enter user-defined coefficients cj on surface(s) sij,
	respectively surface sk. Requires surface type "I" (for gra-
	dient Index) on that surface.

OpTaliX provides a sample subroutine in both FORTRAN and C programming languages. It is found in the directories

\optalix\	usergrn\	Fortran	for FORTRAN
\optalix\	usergrn\	C	for C/C++

with appropriate subdirectories for Lahey/Fujitsu FORTRAN, Intel FORTRAN, Compaq Visual FORTRAN and Microsoft Visual C compilers. Note that the subroutine name must be exactly "usergrn" in small characters and no other name is permitted. The usergrn subroutine can also, if needed, call other subroutines or read data files. The usergrn subroutine that you write in FORTRAN or C must have the following parameters:

usergrn((isur,sdata,x,y,z,wvl,rindx,gx,gy,gz,i\_err)

where:

isur	Current surface number for which the index function and the derivatives are to be evaluated. This is an input parameter which may be used to distinguish between various algorithms on different surfaces. If only one UDG type surface is used, this parameter is normally not needed. See also the note below.
sdata	Data array with 91 elements for passing data between $OpTaliX$ and the usergrn subroutine. The elements of data correspond to the UDG coefficients C1 to C91.
х,у,z	Coordinates at a point along the ray, with z along the optical axis.
wvl	Wavelength, in microns.
rindx	The calculated index of refraction at the point (x,y,z).
gx,gy,gz	A three-element output vector with the x, y, and z components of $\nabla(n)$ at the point
	(x,y,z).
i_err	Error flag. It should be set to 0 if there is no error generated and set to 1 otherwise.

### Notes:

• Only one usergrn subroutine can be linked to *OpTaliX* at one time. Therefore all userdefined gradients in the optical system must use the same usergrn subroutine. However, it is possible to program more than one UDG description with different coefficients in the same usergrn subroutine. The parameter isur designates the surface number currently in use for evaluating index of refraction and derivatives. ! 1

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• If the user-defined gradient has any axial (z) dependence, then the value of "brind" will be negative after a reflector.

### 8.24.14 Default usergrn Subroutine

The default UDG in OpTaliX is the "University of Rochester" type gradient index. The index profile is given by Eq. 8.83 on page 129. The FORTRAN source code of the usergrn subroutine is as follows:

```
subroutine usergrn(isur,sdata,x,y,z,wvl,rindx,gx,gy,gz,i_err)
           Evaluate the function and its derivatives of a user defined GRIN surface
           The function is of the form n\left(x,y,z\right) where \left(x,y,z\right) are the cartesian
           coordinates of a point in the gradient.
           The example GRIN profile is the "University of Rochester" gradient:
           rindx = sdata(1) + sdata(2) * z + sdata(3) * z^2 + sdata(4) * z^3 + sdata(5) * z^4 + z^4 + sdata(5) * z^4 
                           sdata(6)*r^2 + sdata(7)*r^4 + sdata(8)*r^6 + sdata(9)*r^8
           where r^{2} = x^{2} + y^{2}
           Parameters:
           _____
                                : surface number
           isur
                                                                                                                                            (input)
           sdata(91) : Array containing the user-defined GRIN parameters (input)
                                     For example, sdata(1) is the value entered with the
                                     command UCO C1.
           x,y,z
                                 : Coordinates of the current position of the ray with
                                    respect to the origin of the surface
                                                                                                                                           (input)
           wvl
                               : wavelength (in microns)
                                                                                                                                            (input)
                                : The calculated index of refraction at (x,y,z)
           rindx
                                                                                                                                           (output)
           gx,gy,gz
                               : Gradient (derivatives) at coordinates (x,y,z)
                                                                                                                                           (output)
                                     i.e. dn/dx, dn/dy, dn/dz
           i_err
                               : Error flag (0 = no error, 1 = error)
                                                                                                                                            (output)
                                    Note: The error flag must be properly set by the user
           Notes:
           The user will typically substitute his own FORTRAN code for a
           particular surface.
           More than one surface description can be programmed in this subroutine.
           Use the "isur" parameter to distinguish between surfaces and
           determine the interpretation of the coefficients stored in "sdata"
           dll_export usergrn
                                              :: i_err,isur
           integer
           double precision :: x,y,z,gx,gy,gz,rindx,wvl,sdata(91)
           double precision :: rad2,t1,t2,tabl
           i\_err = 0
                                                          University of Rochester Gradient
           rad2 = x \star x + y \star y
! Evaluate index of refraction:
           t1 = z *(z *(z *(z *(z *sdata(5)+sdata(4))+sdata(3))+sdata(2))
           t2 = rad2*(rad2*(rad2*(rad2*sdata(9)+sdata(8))+sdata(7))+sdata(6))
           rindx = sdata(1) + T1 + T2
           if(rindx.lt.1.0d0) then
                 i\_err = 1
                 rindx = 1.0d0
           endif
! Evaluate gradient :
           t1 = rad2*(rad2*(rad2*8.d0*sdata(9) + 6.d0*sdata(8)) + 4.d0*sdata(7))
           tabl = t1 + 2.d0 * sdata(6)
           gx = tabl * x
           gy = tabl * y
           gz = z * (z * (z * 4.d0 * sdata(5) + 3.d0 * sdata(4)) + 2.d0 * sdata(3)) + sdata(2)
```

```
return
end
```

## 8.24.15 Compiling and Linking usergrn

OpTaliX supports the Lahey/Fujitsu FORTRAN, Compaq Visual FORTRAN, Intel FORTRAN and the Microsoft Visual C++ compilers. All supported compilers are 32 bit versions. The 16 bit versions are not supported. All compilers must have version numbers equal or higher as listed below. References to compiler specific instructions are given in the last column.

Manufacturer	Compiler Version	See Section
Lahey Fujitsu	FORTRAN-95, version 5.7 or later	8.31.3
Compaq	Visual FORTRAN, version 6.6 or later	8.31.4
Intel	FORTRAN-95, version 7.1 or later	8.31.4
Microsoft	Visual C/C++, version 5.0 or later	8.31.6

## 8.24.16 GRIN - Coefficients Overview

The parameter C1 to C10 are the coefficients which describe the index *profile* of a gradient index material. To be used in conjunction with the GIC command. The meaning of each profile coefficient depends on the GRIN-type and is defined as follows:

Туре	Equation	C1	C2	C3	C4	C5	C6	C7	C8	C9	C10
SEL	$n_0(\lambda) = c_1 + \frac{c_2}{\lambda^2}$ $\sqrt{A}(\lambda) = k_{11} + \frac{k_{12}}{\lambda^2} + \frac{k_{13}}{\lambda^4}$	$c_1$	<i>c</i> <sub>2</sub>	k <sub>11</sub>	$k_{12}$	k <sub>13</sub>					
GLC	$n(r) = n_0 + n_1 r^2 + n_2 r^4$	$n_0$	$n_1$	$n_2$							
GRT	$n\left(r\right) = n_0 \cdot sech(gr)$	$n_0$	g								
GRC	$n\left(y\right) = n_0 \cdot sech(gy)$	$n_0$	g								
AXG	$n(z) = n_0 + a \cdot z$	$n_0$	a								
								cont	tinued of	on next	page

!

continue	ntinued from previous page										
LPT	$n(z) = n_0 + n_1 \left(\frac{z}{z_m}\right)^1 + $	$z_m$	$n_0$	$n_1$	$n_2$	$n_3$	$n_4$	$n_5$	$n_6$	$n_7$	$n_8$
	$n_2 \left(\frac{z}{z_m}\right)^2 + n_3 \left(\frac{z}{z_m}\right)^3 + \dots + n_{11} \left(\frac{z}{z_m}\right)^{11}$	$n_9$	<i>n</i> <sub>10</sub>	<i>n</i> <sub>11</sub>							
URN	$n(r,z) = n_{00} + n_{01}z + n_{02}z^2 + n_{03}z^4 + n_{04}z^4 + n_{10}r^2$	<i>n</i> <sub>00</sub>	<i>n</i> <sub>01</sub>	n <sub>02</sub>	n <sub>03</sub>	n <sub>04</sub>	<i>n</i> <sub>10</sub>	<i>n</i> <sub>20</sub>	n <sub>30</sub>	$n_{40}$	
	$+ n_{20}r^4 + n_{30}r^6 + n_{40}r^8$										
LUN	$n^2(p) = n_0^2 \left(2 - \frac{p^2}{a^2}\right)$	$n_0$	a	r							
	with $p^2 = x^2 + y^2 + (z - r)^2$										
SPG	$n(p) = n_0 + n_1(r - p) + n_2(r - p)^2 + n_3(r - p)^3 + n_4(r - p)^4$	<i>n</i> <sub>0</sub>	$n_1$	$n_2$	<i>n</i> <sub>3</sub>	$n_4$					
MAX	$n(p) = \frac{n_0}{\left(1 + \frac{p^2}{a^2}\right)}$	$n_0$	a	r							
	with $p^2 = x^2 + y^2 + (z - r)^2$										

# 8.25 Light Pipe, Step Index Fiber

Light pipes and step index fibers are handled in an identical manner. Rays enter a tube (being either solid or hollow) and reflect from the walls an indeterminate number of times until they emerge. Circular and rectangular cross sections are supported. Both end surfaces may have any form (spherical, aspheric, with grating, with surface deformation, etc) and may also be arbitrarily tilted.

Fibers and light pipes are formed by extruded surfaces. The aperture boundary of the entrance surface defines the diameter (= 2\* aperture radius) of the tube and the axial separation to the next surface (the end surface) defines the length of the tube. Thus, the rod conforms to the aperture shape (circular or rectangular) of the entrance surface. In addition, two materials (glasses) must be provided at the entrance surface for core and cladding (use GLA and GL2 commands). The only difference between a light pipe and a step index fiber is in the material for the cladding. In a light pipe, the index of refraction of the cladding is 1, whereas for a step index fiber it is > 1.

The entrance surface of light pipes must have the surface type "P" in addition to the "S" (spherical) or "A" (aspheric) base shape. Example command: sut s3 sp

In a tapered fiber, the cone angle is defined by the semi-diameters of entrance surface and exit surface



Figure 8.34: Light pipe (top) and tapered fiber (bottom).

respectively. In case of rectangular apertures, X- and Y-cross sections of the rod are tapered separately.

Hollow light pipes may be simulated by defining a mirror on the outside walls (not on the end surfaces), which bypasses checking of total internal reflection (TIR). This is accomplished by the command

PMI sij yes no	Pipe Mirror. Enables (yes) or disables (no) reflective properties on
	the outer walls. If enabled, TIR condition will be ignored and rays
	will always reflect at the outer walls.

### Examples:

**Step index** fibers respectively light pipes are completely defined by the following command sequence (supposed, the rod/fiber entrance is at surface 3):

sut	s3	SP	makes surface spherical and defines light pipe respectively fiber
gla	s3	sf6	defines core material
g12	s3	bk7	defines cladding material (gl2 s3 air is a fiber without cladding)
thi	s3	100	length of fiber/pipe is 100mm
cir	s3.	4 2.5	diameter of rod is 5mm (=2*aperture radius)

**Tapered fibers** with circular apertures use the same commands, except that the semi-apertures on entrance surface and exit surface are different:

sut	s3	SP	makes surface spherical and defines fiber/pipe
thi	s3	100	length of fiber/pipe is 100mm
cir	s3	2.5	diameter of entrance aperture is 5mm
cir	s4	1.0	diameter of exit aperture is 2mm. Since the exit diameter differs from
			the entrance diameter, the pipe/fiber is tapered.

The semi cone angle  $\vartheta$  of the tapered fiber in the second example above is then  $\vartheta = tan^{-1}[(2.5 - 1.0)/100].$ 

**Rectangular (tapered) light pipes** have rectangular apertures on both end surfaces. They are defined by the commands:

sut	s3	SP	makes surface spherical and defines fiber/pipe
thi	s3	100	length of fiber/pipe is 100mm
rex	s3	2.5	rectangular aperture, entrance aperture X-diameter is 5mm
rey	s3	2.5	rectangular aperture, entrance aperture Y-diameter is 5mm
rex	s4	1.0	rectangular aperture, exit aperture X-diameter is 2mm
rey	s4	1.0	rectangular aperture, exit aperture Y-diameter is 2mm. Since the exit
			aperture dimensions differ from the entrance aperture dimensions, the
			pipe/fiber is of pyramidal shape.

#### Sheared rectangular light pipe:

The end surface apertures may also be sheared (laterally displaced) at rectangular light pipes. This is accomplished by aperture offsets (see commands ADX, ADY) on the end surfaces. The side walls will automatically be adjusted. Note that shearing of end surface apertures does not shift the optical axis. Aperture offsets are ignored on cylindrical light pipes.

# 8.26 Array Element

The array surface arranges optical elements (surfaces) in a regular grid, i.e. they are repeated many times at specified X/Y locations with respect to the local coordinate of a surface, denoted hereafter as *array cells* or *channel surface*.

The individual lens or surface assemblies may be regarded as *cells* or *channels*. The channel surface encompasses all of the channels in the array. The aperture limits of the array surface are defined by the AMX, AMY parameters. Depending on the aperture dimensions and the cell/channel spacings (ARX, ARY) some channels (array elements) may be truncated. Individual channels are distributed in a uniform grid over the channel surface. The channel centers are located at (local) X/Y coordinates defined by the X-spacing (ARX) and Y-spacing (ARY).



Figure 8.35: Examples of array elements, a) fresnel lens array, b) spherical lens array, c) GRIN rod array. The corresponding example files can be found in the <code>\$i\examples\array</code> directory as <code>sphere-array.otx</code>, <code>fresnel-array.otx</code> and <code>selfoc-array.otx</code>.

Array surfaces are defined by the surface type qualifier "R" in addition to any other qualifier describing the shape of the surface (e.g. "S" or "A") to be repeated.

А	RR sij x_s	spacing y_spacing x_offset y_offset max_x max_y				
	Convert surface(s) sij to an array, using a regular grid pattern of channels.					
	The channel coo	ordinates (centerlines) are determined by				
	x_spacing	Grid spacing in X-direction between				
		channel centers.				
	Y_spacing	Grid spacing in Y-direction between				
		channel centers.				
	x_offset	Offset of center channel from surface				
		vertex in X-direction.				
	y_offset	Offset of center channel from surface				
		vertex in Y-direction.				
	max_x	$\pm$ limit for grid in X-direction				
	max_y	$\pm$ limit for grid in Y-direction				
	-					

	Array hexagonal arrangement.
ARH sk sij Y N	ARH sk Y : hexagonal cells arrangement (Fig. 8.37),
	ARH sk N : cells arranged in rectangular grid (Fig. 8.36).
ARX sk sij x_spacing	X-spacing of array channels.
ARY sk sij Y_spacing	Y-spacing of array channels.
ARXO sk sij X_offset	X-offset of entity of array channels with respect to local surface
	coordinate system.
ARYO sk sij Y_offset	Y-offset of entity of array channels with respect to local surface
	coordinate system.
AMX sk sij max_x	$\pm$ limit for grid in X-direction
AMY sk sij max_y	$\pm$ limit for grid in Y-direction
AADE sk sij	$\alpha$ -tilt angle (in degree) of each array cell.
angle_deg	
ABDE sk sij	$\beta$ -tilt angle (in degree) of each array cell.
angle_deg	
ACDE sk sij	$\gamma$ -tilt angle (in degree) of each array cell.
angle_deg	

Array properties can be combined with any type of surface, i.e. spherical, aspheric, Fresnel, GRIN and so on. For example, the following commands define various valid combinations of array surfaces:

sut	s1	SR	Defines surface type for an array of spherical surfaces
sut	s1	AR	Defines surface type for an array of aspheric surfaces
sut	s1	SFR	Defines surface type for an array of Fresnel surfaces with spherical base
			curvature
sut	s1	SIR	Defines surface type for an array of GRIN surfaces with spherical base
			curvature

There can be as many arrays as are surfaces in the optical system. Lens arrays, which span more than one surface (i.e. elements) can be generated by repeating the array parameters from previous surfaces. The apertures of the array channels are defined by the surface apertures (see CIR, REX, REY, ELX, ELY commands).

If both, x\_spacing and y\_spacing are zero on a given surface, the array property is ignored and the lens behaves like a continuous (non-array) surface.



Figure 8.36: Definition of array parameter shown for a square regular grid. The dashed lines indicate the vertex of the base surface.

#### **Restrictions:**

- 1. Array parameters may not be zoomed. Parameters of the channel surface such as curvature, thickness, etc may be zoomed.
- 2. Array parameters may not be used in optimization.

#### **Example:**

An array of spherical channel surfaces as shown in Fig. 8.35(b) is best created when starting from a plano-convex lens. The first surface of the lens is converted to an array by

arr s1 5 5 0 0 15 15

where the spacings of the channel centerlines are 5mm in X- and Y-direction. The qualifier "R" is correspondingly added to the surface type without requiring user interaction. The X- and Y-offsets are zero. This aligns the center channel on the vertex of the base surface. The extent of the array is given by the  $\pm$  data pair (15 15). We may also enter the ARR command by discrete commands:

sut s1 sr arx s1 5 ary s1 5 arxo s1 0 aryo s1 0 amx s1 15 amy s1 15

Next we will reduce the radius of curvature of surface 1 to pronounce the effect.



Figure 8.37: Hexagonal arrangement of array cells. All odd numbered columns are shifted (staggered) in Y-direction by 0.5\*ARY. Optimal packaging of cells is then accomplished with ARX =  $\cos(30^\circ)$ \*ARY = 0.866\*ARY.

#### rdy s1 3

and will also define a fan of 31 rays along the Y-direction in order to better visualize refraction of rays in the lens layout plot (see also VIE command).

set fan y 31

The output should be as shown in Fig. 8.35(b).

## 8.27 Radial Spline Deformation Surfaces

The radial spline deformation surface is rotationally symmetric about the vertex of the base surface. The radial spline is defined by deformation points in radial direction, starting from the vertex to the outer rim of the surface. Each deformation point is described by a pair of two values, the radial distance (SPLR) from the vertex and the deformation value (SPLZ) perpendicular to the base surface. The base surface can be any of the surface types available in OpTaliX, for example a sphere or asphere. Since the spline function is added to the base surface, the surface type (SUT) must be composed of two letters, e.g.

SC = spherical base surface + spline AC = aspherical base surface + spline

Up to 20 radial deformation points are supported per surface. There may be as many spline surfaces as are surfaces in the current system. The deformation points are then fitted by a "Spline" interpolation method to obtain a continuous radial function across the surface. It should be noted that the deformation points are simulated exactly while all intermediate coordinates may exhibit "overshoot-ing" effects which are generally not desired. Since spline interpolation attempts to generate "smooth" curves (i.e. first and second derivative of two adjacent segments match), there is no direct control

of the surface slope. This behaviour is inherent to the Spline fitting method and does not constitute an implementation fault. A finer (smaller) sampling interval should be chosen in such cases. It is also good practice to provide additional sampling points outside the active area (if available) to avoid boundary effects. In some cases, when the spline deformation is very steep, a ray passing the exact surface vertex at exact normal incidence of the local surface may be deviated. This is also a boundary effect which may be reduced (or eliminated in most cases) by adding an extra sampling point close to the vertex point of the surface. This forces a zero slope at this point.

SPLN sij	Number of (radial) spline deformation points at surface(s)
n_spline_points	sij
	Radial distance from the vertex of the surface(s) sij. The
	radial distances are measured along the vertex tangent plane.
SDID si i si i	Example:
rad digt1	splr s3 c15 0 2 4 7 13
rad dist n	where the deformation points are located at 0,2,4,7 and 13mm
	from the surface vertex.
SPLZ sij cij def_1	Deformation from the base surface, measured perpendicular to
def_2 def_n	the normal of the base surface. Example: splz s3 c15
	0.0 0.001 -0.002 0.003 -0.004
	Load Spline deformations from file "file_spec". A detailed
	description of the radial Spline file format is given in section
SPL sij file	32.5.
file_spec	Example:
	spl s4 file c:/temp/spline_def.dat

### Example:

We will apply a periodic deformation of roughly sinusoidal shape for easy visualization of the effects. First, we will enter the data manually in the command line and later on will learn about importing (loading) the spline deformation stored in a file. Assuming 6 sampling points, the command sequence is (without entering the exclamation mark and the text right to it)

```
      spln 6
      ! define number of sample points

      splr s1 c1..6 0 0.001 10 20 30 40
      ! define the radial distances

      splz s1 c1..6 0 0 .001 -.001 .001 -.001
      ! define the deformation
```

Note the second sampling point, which has been set very close to the first sampling point. This forces a zero slope at the vertex in the spline interpolation.

Alternatively, we could edit the data in a separate text (ASCII) editor outside of OpTaliX and store it in a file. It is then loaded with a single command. Using the demonstration example above, the file would look like (with comments included)

```
! Spline deformation file
0 0
0.001 0 ! this is an extra data point
10 0.001
20 -0.001
30 0.001
40 -0.001
! end of file
```

See also section 32.5 for a detailed description of the radial Spline file format. The file is loaded with the command SPL s1 file 'c:\optalix\my-spline-data.spl'. Path and file-name must be adjusted accordingly.

# 8.28 Two-Dimensional Interferometric Deformation on Surfaces

Interferometric deformations are specified as two-dimensional gridded data. Using this method, nonrotationally symmetric deformations can be modelled. Typically, such data is obtained from interferometric measurements of lens surfaces or complete optical systems or from external programs that generate appropriate data files. The surface type (SUT) must have the qualifier "W" in order to make 2-dimensional deformation/apodization data active.

The data in an interferogram file can represent either surface deformation, wavefront perturbation data or intensity apodization data:

- Surface deformation data is added to whatever surface shape is defined with the lens. Deformation data is always measured normal to the nominal surface. During ray tracing, both ray aberrations and wave aberrations will be properly modified. Surface deformation data are always associated with refractive or reflective surfaces, they have no effect on dummy surfaces (same medium on both sides of a surface).
- Wavefront perturbation data modify the ray deviations and optical path difference (OPD) but has no effect on surface shape, even though it is associated with a (refracting/reflecting) surface.
- **Intensity apodization data** modify the transmission characteristics of an optical system but do not alter surface shape and ray directions.

Interferometric deformations can be scaled in deformation (ISF) and its origin can be placed at a particular X,Y location on the surface (INX and INY commands).

A file interface is provided that allows reading (importing) two-dimensional data sets. This data (surface deformation, wavefront perturbation or filter) is then assigned to a surface.

INT sk file int_file_name	Assign surface deformation data given in the file int_file_name to surface sk. No particular exten- sion of the file name is required, however, ".int" is rec- ommended. The file format must obey a specific struc- ture, which is specified in section 32.11.
ORB sk file orb_file_name	This command is functionally equivalent to the "INT" command above, except that it expects surface deformation data in a form provided by the "Orbscan II" topography system from Bausch & Lomb used in surgical treatments of the human eye. The data must have been exported in cartesian form (gridded data) using the "Recorder" option. The surface deformation data in the file orb_file_name is then attached to surface sk.
	continued on next page

continued from previous page		
ISF sij scale_factor	Scales the measured deformation by a specified scale factor. For example, a scale factor 0.5 is often used for scaling of surface data obtained in a double-pass interferometric setup. A scaling factor -1.0 also allows flipping the deformation data from "bump" to "dent".	
INX sk x_offset	X-coordinate on surface sk where the center of the de- formation data is placed.	
INY sk x_offset	Y-coordinate on surface sk where the center of the de- formation data is placed.	
IRX sk x_extension	Physical extension of the deformation array in X-direction on surface sk. Extension is meant as $\pm$ value from the center of the deformation data.	
IRY sk y_extension	Physical extension of the deformation array in Y-direction on surface sk. Extension is meant as $\pm$ value from the center of the deformation data.	
PLO INT [sk]	Plots two-dimensional deformation assigned to surface sk. See also sect. 8.28.8.	
RAW2INT file raw_file	Convert two-dimensional gridded data in "raw" for- mat to INT format. This is a utility command which is useful when only "raw" data are available. The file raw_file must be provided in ASCII format with full path specification. The parameter "file" is mandatory. The data in the RAW format may be sep- arated by blank characters, comma, tabs or by quote characters ". One line in the ASCII file corresponds to one row in the data grid. Thus, there are as many lines in the the file as are rows in the data array. The file must not contain any header or comment lines. The array size is extracted from the data itself. <b>Example:</b> raw2int file c:\mydata.txt The converted data are then written in a separate file in the same directory with the extension .int ap- pended. From the example above, the output (con- verted) file is then c:\mydata.txt.int	

## 8.28.1 Saving Deformation Data

Deformation data associated to surfaces in the current optical system can be saved in two variants:

a) The deformation data are kept in the original file and only a "link" to the file containing the data is saved with the prescription data. This method allows small prescription files, however, an absolute path is stored. However, absolute paths cannot be updated when your computer configuration changes. For example, if you change the location of the deformation file (move

it) or send your prescription file to anybody else (via Internet/Intranet) who most likely has a different directory structure on his computer, OpTaliX will not be able to find the deformation file. Only in cases where you can relay on a stable and consistent file structure, saving links is recommended.

b) The second option, which is independent on file structure, saves the deformation data as an integral part of the prescription data. Large file sizes may result, depending on the number of surfaces that have deformations associated and on the array sizes of the deformation data itself.

Saving deformation data is controlled by from the command line by

	Save interferometric deformation, wavefront or filter data as link
ILN Yes No	to a file. On saving or restoring an optical system, the data are
	retrieved from the original file (ILN YES) or are stored along
	with the description data (ILN NO). There are specific advan-
	tages/disadvantages in choosing either method:
	ILN YES : Only stores a link to the file containing the data (INT,
	BMP, PCX or PNG file). On restoring the optical system, the file
	must exist, i.e. accessible by path and file name. Moving files may
	result in loss of data due to inaccessible files.
	ILN NO: Saves all data with the prescription data. The corre-
	sponding $OpTaliX$ file may become VERY large, depending on
	the amount of data involved in describing the perturbation or filter
	characteristics. This way, perturbation data will always be available,
	however, it cannot be changed except by reloading new data.

or from the configuration dialog invoked from the main menu by Edit - > Configuration Data. In the *General* tab, check the option "*Store 2-dim deformation with prescription data*", as shown in Fig. 8.38.

Optical System Configuration	
Aperture Fields Wavelengths General Astigmatic Object	
Afocal (in image space)	
<ul> <li>Spectrometer Mode (overlays Fan and Spot aberrations irrespective of chief ray coordinate)</li> </ul>	
Extend GRADIUM profile beyond material limits.	
Store 2-dim deformation data with prescription data	
Include Transmission	
✓ Include Polarization	
Maximum Frequency (MFR) : 50.000 Update Graphics: never	

Figure 8.38: Option for saving interferometric deformation data, wavefront or filter data. Check if data are to be saved with prescription data, leave unchecked if data are maintained in separate file, accessed by a link.

**Caution:** Once 2-dimensional deformation data are stored with the prescription data and the appropriate check box in the configuration dialog has been checked, it is not recommended to uncheck it. If unchecked, the program does not know where to store the deformation data, since it cannot create the original files, and the data will be lost. That is, the program provides two methods of handling and storing deformation data, however, the storing method should not be changed after a selection has been made.

### 8.28.2 Sign Conventions

A positive deformation in the data file(s) is in the direction of the local Z-axis for the surface, regardless of the direction of light. Thus, the physical meaning depends on which side of an optical element is considered. For a singlet lens, for example, a positive deformation on the first surface is a concave increment ("dent") to the surface while a positive deformation on the second ("rear") surface is a convex increment ("bump") to the surface.



Figure 8.39: Sign convention for two-dimensional deformations on surfaces.

It is generally a good idea to test the correct orientation of coordinate axes (X,Y) of deformation data with marked pieces. A plot of the deformation data as shown in Fig. 8.40 is helpful to visualize the data in the OpTaliX coordinate system. This plot is generated by the command (on the example of surface 3)

plo int s3 or from the menu: *Display* -> *Show 2-dim. Surface Deformation* 

## 8.28.3 Interferometric Deformation Data

Surface deformations obtained from interferometric measurements or from other external programs (e.g. NASTRAN deformations) are read in by the INT command. The file format is identical to the Code V INT-files and is specified in section 32.11.

Due to the inherent structure of Code-V INT files, no provision for specifying the lateral X- and Yextensions of the data, respectively the coordinates of the X/Y sample points, is foreseen. Thus, the connection of the unit length of the file data to the physical length on the surface must be specified separately. To control the correct X/Y-extensions on a specific surface use the PLO INT command.

In OpTaliX mapping of the file data to the surface aperture is queried at the time of loading/assigning deformation data as shown in Fig. 8.41.

## 8.28.4 Wavefront Perturbations

Wavefront perturbation data must be provided in the INT file-format (see section 32.11 on page 523) as defined in Code V. This means that Code V INT files can be directly read in and associated to surfaces without modification.


Figure 8.40: Plot of two-dimensional surface deformation in the OpTaliX coordinate system. The deformation is always shown in the direction of the positive Z-axis. For systems having no mirrors or tilted components, the positive Z-direction is identical to the direction of light (from left to right in the lens layout plot).

Wavefront perturbations modify the ray directions and the optical path difference (OPD) but there is no effect on surface shape, even though it is associated to a surface. Wavefront perturbations are usually placed on dummy surfaces. Wavefront perturbation data can be viewed using the PLO INT command.

## 8.28.5 Surface Intensity Apodization (Intensity Filter)

Intensity apodization data are read in from an INT-file or a bitmap file (BMP, PCX or PNG) and are associated to a specific surface. Surface based apodization only modifies the intensity transmission along a ray path and thus can be understood as a spatial intensity filter. There is no effect on surface shape and direction of rays. By default, rays are not blocked, except in regions where data is missing (see sect. 8.28.7). In addition, rays can be blocked in regions of zero intensity if the IBZ attribute is assigned to a filter (sect. 8.28.7).

Intensity apodization can be associated to any surface (except object and image surface), however, they are typically associated to dummy surfaces. The effect of the apodization on the beam profile depends upon the region of the surface that is hit by the beam.

Apodization filter data in INT-files or BMP/PCX/PNG files are transmission and can have any value grater than 0. See a detailed description of the INT file format in section 32.11. Apodization filters can also be defined in a bitmap file (BMP, PCX or PNG) in which transmission is grey-coded in grey levels between 0 (no transmission) and 255 (full transmission = 1.0).

Apodization filters can be placed on surfaces with X- and Y-offsets using the INX and INY commands. Inversion and scaling of intensity data is not possible. Use the PLO INT command to control correct placement and scaling of apodization data on surfaces. The effect of intensity apodization on system transmittance can be plotted by the pupil intensity map (PMA) option as described in section 14.1.9.

It is not required to activate transmission analysis (TRA yes|no) or polarization analysis (POL yes|no) to see the effects of intensity apodization filters on performance. Once attached to a surface,

📢 Interferometric Deformation
Attach interferometric deformation to surface:
Surface 1
Deformation Scale Factor, ISF: 1.0000
Deformation Offsets: INX: 0.000 INY: 0.000
Match data to free aperture dimensions
Extension of measured data, X: 2.500 Y: 2.500
Help Cancel OK

Figure 8.41: Assigning two-dimensional deformations from Code V compatible INT files to surfaces and specifying scaling factor and X/Y offsets. The connection of the unit length (maximum array size) to the physical extension on the surface can be accomplished by matching the data to the clear surface aperture (default) or by explicitly specifying X/Y extensions of the interferogram data.

intensity apodization filters are always active.

#### 8.28.6 Deformations from Orbscan II Topography System

Surface deformation data obtained from the "Orbscan II" topography system from Bausch & Lomb are assigned to surfaces using the ORB command. It is functionally equivalent to the INT command, except that a different file format is expected.

The Orbscan II data must be provided in cartesian form (gridded data) using the "Recorder" option (see the Orbscan manual). This option writes a readable ASCII file. Orbscan topographic data can be read in and assigned to optical surfaces from the command line or by selecting menus. For example, importing Orbscan II deformation data is accomplished in the command line by

```
orb s3 file c:\temp\def_data.txt
```

The file may have any extension. Note the use of the expression "file" in the command. It is required to identify the subsequent string as a path and file specification. Using menu items, the same file is assigned to surface 3 by clicking

#### File -> Import -> Orbscan Map Data

Select the file containing the deformation data from the file selection box. The surface association is performed in a subsequent dialog box as shown in Fig. 8.42. It also allows definition of the (interferogram) scaling factor ISF, which is used to change the sign of the deformation data, as well as X- and Y-offsets (INX, INY) where the deformation is placed on the surface.

Orbscan map data are defined and stored in a left-handed coordinate system. Since the coordinate system used in OpTaliX is also left-handed, no special precautions such as inverting or mirroring data is required. In particular, ISF should be +1.0.

(🐝 Ir	mport Orbscan II Map Data			_ 🗆 ×
	Attach Orbscan II Map Data to surfa	ice:		
	Surface 1			
	Deformation Scale Factor, ISF:	1.0000		
	Deformation Offsets: INX:	0.0000	INY:	0.0000
	Match data to free aperture dim	ensions		
	Extension of measured data, $\times$ :	0.0000	Y:	0.0000
	Help Cancel		ОК	

Figure 8.42: Assigning Orbscan map data (two-dimensional deformations) to surfaces and specifying scaling factor and X/Y offsets. The lateral X/Y extensions are greyed out, because these are explicitly provided with Orbscan files and need not specified.

### 8.28.7 Behaviour of Rays in Regions of No Data

Interferogram or filter data can have regions of missing data. Possible reasons may be clipping by the edge or obscuration of the piece being tested, noise or too weak signal in the interferometer detector, or other reasons. Missing data are indicated in the files according to the value associated with the NDA file entry.

Rays which hit "no data" regions will be blocked, irrespectively whether the surface aperture is checked (fixed aperture) or not.

Optionally rays can also be blocked on surfaces with intensity filters if the intensity reaches zero. The IBZ flag controls behaviour of rays in such regions:

	Block rays in regions of zero intensity. This option is <i>only</i> applicable
	on surfaces with intensity filters. If this flag is set (IBZ sk YES),
	rays hitting a region where the intensity approaches zero ( $< 0.001$ )
	are blocked. Specify IBZ sk NO to let rays pass irrespective of the
	intensity imposed by the filter.
IBZ sıj sk	
Yes No	The IBZ option is particularly useful to model very complex aperture
	shapes. Any arbitrary shape provided in an INT-file or a bitmap file
	(BMP,PCX,PNG) may be attached as an intensity filter. IBZ YES
	on that surface will then define the complex aperture as all rays at
	zero intensity will be blocked.

#### 8.28.8 Display Interferometric Deformation

Interferometric deformations attached to a surface can be viewed by the PLO INT command:

PLO INT sk [?]	Plot interferometric deformation attached to a surface. The question
	mark (optional) invokes a dialog box for editing plot parameters.

A sample plot of an interferometric deformation and the associated surface aperture is shown in Fig. 8.43 (page 148). This plot allows mapping of the interferogram file data to the surface aperture. Notice that the interferogram dimensions are queried at the time of loading/assigning deformation data. However, interferogram dimensions can be changed by the IRX, IRY commands.



Figure 8.43: Display interferogram deformation on a surface. The surface aperture is shown in red colour which allows a direct comparison with the measured interferogram dimensions.

Interferometric deformations can be plotted in four styles, wire-grid plot, gray-scale plot, false-colour plot and as X/Y-sections. Currently, the plot style can only be defined within the option dialog box (i.e. PLO INT ?).

## 8.29 Zernike Surface

The Zernike surface is defined by the surface type "Z" which may be added to any other base surface (e.g. spherical, aspherical, toroidal, etc). Zernike surfaces are always defined in terms of "Finge Zernike polynomials". Zernike surfaces may be defined as surface or phase deformation:

- Zernike **surface** deformation: Defines a deformation of the surface, i.e. direction and optical path along a ray are altered by the law of refraction. The Zernike surface deformation is preferably applied to surfaces with an air/glass or glass/air interface.
- Zernike **phase** deformation: Introduces an additional phase component to the optical path (wavefront). The direction of rays is modified such that rays are always perpendicular to the phase additive. Zernike phase surfaces must be defined on surfaces with the same medium on both sides of the surface (preferably AIR/AIR interfaces).

#### **Command Overview:**

ZRN [sii sk]	Define Zernike deformation on surface (SUR), or as
SURIPHA	phase/wavefront perturbation (PHA) at surface(s) si i The
501(1111	Zernika surface deformation is preferably applied to surfaces
	with sin/sloss respectively sloss/sin interfaces the Zernike
	with an/glass, respectively glass/air interfaces, the Zernike
	phase surface should only be applied to air/air surfaces (i.e.
	dummy surfaces).
	Define Zernike type, i.e. the sequence of the Zernike coefficients.
	Currently, the following Zernike definitions (types) are supported:
ZTYP ZFR ZFE ZRN	ZFR : Fringe Zernike polynomials
[sij sk]	ZFE : Extended Fringe Zernike polynomials
	ZRN : Standard Zernike Polynomials
	Code V compatibility command to the ZTYP command (as above)
	Sets the following Zernike definitions (types):
SDS 7FD 7FF 7DN	ZER : Eringe Zernike polynomials
	ZER : Extended Eringe Zemike polynomials
	ZFE. Extended Finige Zennike polynomials
	ZRN : Standard Zernike Polynomials
ZRN [sij sk] cij	Set Zernike coefficient ci i at surface(s) si i
SCO [sij sk] cij	
	Load Zernike deformation coefficients from file f_name and at-
	tach it to a specific surface sk or a range of surfaces sij. A
ZRN SIJ SK FIL	description of the Zernike coefficients file format is given in sec-
f_name	tion 32.4.
	Fit Zernike polynomials to wavefront aberration at field fi at the
	reference wavelength. Make sure to have appropriate Zernike co-
ZRN WAV [fi]	efficients on wavefront activated (see ZWACT command below)
	See also the WZRN command to retrieve Zernike coefficients fit-
	ted to the wavefront
PLO ZRN si	Plot Zernike-wave based on Zernike coefficients associated to
	surface si
FDI 7DN ci	Onans a dialog how to add Zarnika coefficients associated to
LUI AUN SI	opens a dialog box to cuit Zernike coefficients associated to
INK [S1] SK] radius	Connects the unit circle of Zernike data to a physical aper-
	ture on the surface(s) $s_1$ $i \mid s_k$ The entered value is the
	radius on that surface(s) The default value for TND is the corrit
	liamaten of the surface clean anester. Note: If the clean of
	diameter of the surface clear aperture. <b>Note:</b> If the given value
	of radius scales the Zernike deformation to a smaller value than
	the actual semi-aperture, the data outside the INR radius will
	be extrapolated, leading to false results! This case must be
	avoided.
	continued on next page

continued from previous page				
ZACT sij sk cij act1 act2	Activate/deactivate Zernike coefficients on a particular surface (or range of surfaces). Activating a coefficient means that it will be used in the performance analysis. "act" is an integer number of 0 or 1, where 0 deactivates a coefficient and 1 activates it. In ab- 			
ZWACT cij act1 [act2]	Activate/deactivate Zernike coefficients used for wavefront fitting. Activating coefficients means that they will be used for fitting the wavefront. "act" is an integer number of 0 or 1, where 0 de- activates a coefficient and 1 activates it. In absence of a coeffi- cients specifier "c", a sequence of integer values is expected (see third example below. A surface qualifier is not required, since the ZWACT switches always apply to the wavefront Zernike coeffi- cients. Examples: zwact c1 1 ! activates Zernike coeffi- cient 1 to be used for wave- front fitting, zwact c15 1 ! activates Zernike coeffi- cients no. 1 to 5 for wave- front fitting, zwact 1 0 1 0 1 ! activates coefficients no. 1,3 and 5, deactivates coeffi- cients no. 2 and 4. Alternatively, wavefront coefficients may be activated/deactivated in the Zernike spreadsheet editor, which is invoked by the com- mand EDI ZRN (see above). Use the command WAV ZRN to actually fit the coefficients to the wavefront aberration at a par- ticular field. For the definition of Zernike coefficients see sect. 8.29.2).			
WZRN Cij	Set Zernike coefficients cij of wavefront. Fit Zernike coefficients to the actual wavefront at a specific field using the ZRN WAV command. (see above) and subsequently edit them by the EDI ZRN command.			
	continued on next page			

continued from previous page	
WZRN Ck fk	In macros or from the commandline, retrieve a specific wavefront Zernike coefficient, where ck is the k <sup>th</sup> coefficient, and fk is field k. Example: eva [wzrn c3 f1]

#### Example 1:

Typical surface irregularities caused by fabrication errors can be simulated by adding Zernike deformations to particular surfaces. A likely effect in "synchro-speed" generation of spherical surfaces can be modelled with good approximation using only one Fringe Zernike term, Z9, as shown in Fig. 8.44. We assume a measured irregularity  $\tau = 0.5 wavesPV$  at 633nm on a surface exhibiting only this defect. Since in the unit circle  $-0.5 < Z_9 < 1.0$ , the PV value of  $Z_9$  in the unit circle is 1.5, the coefficient  $Z_9$  calculates to

$$Z_9 = \frac{\tau \cdot \lambda_{633}}{PV_{unit-circ}} = \frac{0.5 \cdot 0.000633}{1.5} = 2.11 \cdot E^{-4}$$
(8.87)

 $\lambda_{633}$  is the interferometer wavelength (633nm). This deformation is entered by the following commands (without typing the exclamation mark and the text right to it):

SUT s2 SZ! surface type is spherical + ZernikeZRN s2 c9 2.11e-4! enters Zernike coefficient Z9 at surface 2

Alternatively, we may enter the coefficients in the Zernike spreadsheet editor, which is invoked by the EDI ZRN command. Find a more detailed explanation of the Zernike spreadsheet editor in section 8.29.1, page 152. The surface type can be changed in the surface spreadsheet editor, (use command EDI SUR, if not already open).



Figure 8.44: Fringe Zernike deformation, using only coefficient 9.

#### Example 2:

Fitting Zernike polynomials to the actual wavefront aberration at a particular field is accomplished with the ZRN WAV command. Suppose, we want to see the Zernike terms at field 2, we must first specify, which coefficients are to be included (activated) in the fitting process. Subsequently, fitting can be performed. Both operations are done, for example, by the commands

ZWACT	0	1	1	1	1	1	1	1	! activate Fringe Zernike coefficients 2-8 for wave-
									front fitting. Coefficients 1 and 9-36 are excluded
									from fitting.
ZRN W	AV	f2							! Perform Fringe Zernike fitting of system wavefront
									at field 2.

and obtain the following output of the fitted Fringe Zernike coefficients at field 2 (the reference wavelength number is 2):

```
Zernike polynomial fit of wavefront at field 2 colour 2
          coefficient
                         coefficient
                                       Description of Fringe Zernike Coeff.
      (unit = micron) (unit = wave)
                        -1.39053
  2
        -0.817072827
                                         Y-Tilt
  3
          1.184744104
                             2.01624
                                        Defocus
         -1.401898817
                             -2.38580 Astigmatism 3rd Order, 0 and 90 deg.
  4
         0.00000000
                             0.00000 Astigmatism 3rd Order, +/- 45 deg.
  5
          0.00000001
  6
                             0.00000 X-Coma and Tilt, 3rd Order
                             -3.73022 Y-Coma and Tilt, 3rd Order
2.46817 Spherical and Focus, 3rd Order
  7
         -2.191878576
  8
          1.450299352
```

#### 8.29.1 Zernike Spreadsheet Editor

Editing of Zernike coefficients can be performed in a more convenient manner via the Zernike spreadsheet editor (see Fig. 8.29.1). It is started from the command line by EDI ZRN and allows input of Zernike deformation coefficients at surfaces as well as fitting of the wavefront aberration. Any surface in the optical system (except the object and image surface) may be selected. If "wavefront" is selected, the Zernike coefficients relate to the wavefront aberration in the exit pupil. For this case, it does not make much sense to enter coefficients (although it is possible), but this option is merely used to fit a Zernike polynomial to the existing wavefront. Select (activate) in the second column, which coefficients shall be included in the fit.

Zernike coefficients may be loaded from a file or stored into a file. The latter is particularly useful for fitted wavefront aberrations.

#### 8.29.2 Definition of Zernike Polynomials

Zernike polynomials are circle polynomials in radius and azimuth. They are favoured in representing wavefront because they are orthogonal and normable within the unit circle. This implies that each term is independent from all others. Therefore, neither the inclusion or exclusion of a given term will affect the values of the other terms. This is strictly true only for continuous data, but it is approximately true for data that is uniformly spaced over a circular aperture. The Zernike polynomials have the general form

$$Z_n^m(r,\phi) = R_n^m(r) \left[\cos m\phi + \sin m\phi\right]$$
(8.88)

where r and  $\phi$  are polar coordinates within the unit circle. Typically, wavefront data are represented in the pupil of an optical system in cartesian pupil coordinates  $x_p, y_p$ . The relationship between  $[r, \phi]$ and  $x_p, y_p$  is

$x_p$	=	$r\cos\phi$	(8.89)
-------	---	-------------	--------

$y_p = r \sin \phi$	(8.90)
---------------------	--------

Zernike Loemcients					
Surface :		Coefficient	On	Var	Description
1 💌	1	0.000000			Offset
	2	0.000000			X-Tilt
Deformation type	3	0.000000			Y-Tilt
Surface	4	0.1000000E-03	•		Defocus
Phase	5	-0.3650000E-03	•		Astigmatism 3rd Order, 0 and 90 deg.
	6	0.000000			Astigmatism 3rd Order, +/- 45 deg.
1 1 1 1 1 1	7	0.5000000			X-Coma and Tilt, 3rd Order
Load coerrs from file	8	0.5873000E-04	•		Y-Coma and Tilt, 3rd Order
Save coeffs to file	9	0.00000			Spherical and Focus, 3rd Order
Et bedenne fan it	10	0.00000			Triangular-X, 5th Order
Fit Wavemont	11	0.00000			Triangular-Y, 5th Order
Show Zernike	12	0.00000			Astigmatism, 5th Order
Deformation	13	0.000000			Astigmatism, 5th Order
	14	0.00000			Coma, 5th Order
Help Close		0.000000	_		

activate / deactivate coefficients

coefficient is variable in optimization

Figure 8.45: Editing of Zernike coefficients at surfaces, respectively fitting of wavefront aberration.

We shall be concerned in the following treatment with the Fringe ZERNIKE polynomials, the extended Fringe Zernike polynomials and the standard Zenike polynomials according to Born and Wolf [4].

#### 8.29.3 Fringe Zernike Polynomial Terms (ZFR)

The Fringe Zernike polynomial set is limited to 36 terms with a higher order radial term ( $49^{th}$  term of the **extended** Fringe coefficients) appended as the  $37^{th}$  term.

Term	n	m	FRINGE-Zernike-Polynomial	Meaning
1	0	0	1	Offset
2	1	1	$Rcos(\phi)$	X-Tilt
3	1	1	$Rsin(\phi)$	Y-Tilt
4	2	0	$2R^2 - 1$	Defocus
5	2	2	$R^2 cos(2\phi)$	Astigmatism 3 <sup>rd</sup> order
				at $\phi = 0$ or $90^{\circ}$
6	2	2	$R^2 sin(2\phi)$	Astigmatism 3 <sup>rd</sup> order
				at $\phi = \pm 45^{\circ}$
7	3	1	$(3R^3 - 2R)cos(\phi)$	X-Coma and tilt, $3^{rd}$ or-
				der
8	3	1	$(3R^3 - 2R)sin(\phi)$	Y-Coma and tilt, $3^{rd}$ order
9	4	0	$6R^4 - 6R^2 + 1$	Spherical and focus, 3 <sup>rd</sup>
				order
				continued on next page

Table 8.34: Fringe Zernike Polynomials (ZFR)

continued from previous page				
10	3	3	$R^3 cos(3\phi)$	Triangular-X, 5 <sup>th</sup> order
11	3	3	$R^3 sin(3\phi)$	Triangular-Y, 5 <sup>th</sup> order
12	4	2	$(4R^4 - 3R^2)\cos(2\phi)$	Astigmatism, 5 <sup>th</sup> order
13	4	2	$(4R^4 - 3R^2)sin(2\phi)$	Astigmatism, 5 <sup>th</sup> order
14	5	1	$(10R^5 - 12R^3 + 3R)cos(\phi)$	Coma, 5 <sup>th</sup> order
15	5	1	$(10R^5 - 12R^3 + 3R)sin(\phi)$	Coma, 5 <sup>th</sup> order
16	6	0	$20R^6 - 30R^4 + 12R^2 - 1$	Spherical, $5^{th}$ order
17	4	4	$R^4 cos(4\phi)$	Quadratic-X, 7 <sup>th</sup> order
18	4	4	$R^4 sin(4\phi)$	Quadratic-Y, 7 <sup>th</sup> order
19	5	3	$(5R^5 - 4R^3)cos(3\phi)$	Triangular, 7 <sup>th</sup> order
20	5	3	$(5R^5 - 4R^3)sin(3\phi)$	Triangular, 7 <sup>th</sup> order
21	6	2	$(15R^6 - 20R^4 + 6R^2)\cos(2\phi)$	Astigmatism, 7 <sup>th</sup> order
22	6	2	$(15R^6 - 20R^4 + 6R^2)sin(2\phi)$	Astigmatism, 7 <sup>th</sup> order
23	7	1	$(35R^7 - 60R^5 + 30R^3 - 4R)cos(\phi)$	Coma, 7 <sup>th</sup> order
24	7	1	$(35R^7 - 60R^5 + 30R^3 - 4R)sin(\phi)$	Coma, 7 <sup>th</sup> order
25	8	0	$70R^8 - 140R^6 + 90R^4 - 20R^2 + 1$	Spherical, 7 <sup>th</sup> order
26	5	5	$R^5 cos (5\phi)$	5-fold, 9 <sup>th</sup> order
27	5	5	$R^5sin(5\phi)$	5-fold, 9 <sup>th</sup> order
28	6	4	$(6R^6 - 5R^4)\cos(4\phi)$	Quadratic, 9 <sup>th</sup> order
29	6	4	$(6R^6 - 5R^4) \sin(4\phi)$	Quadratic, 9 <sup>th</sup> order
30	7	3	$(21R^7 - 30R^5 + 10R^3)\cos(3\phi)$	Triangular, 9 <sup>th</sup> order
31	7	3	$(21R^7 - 30R^5 + 10R^3) \sin(3\phi)$	Triangular, $9^{th}$ order
32	8	2	$\left(56R^8 - 105R^6 + 60R^4 - 10R^2\right)\cos(2\phi)$	Astigmatism, 9 <sup>th</sup> order
33	8	2	$(56R^8 - 105R^6 + 60R^4 - 10R^2)\sin(2\phi)$	Astigmatism, 9 <sup>th</sup> order
34	9	1	$\left(126R^9 - 280R^7 + 210R^5 - 60R^3 + 5R\right)\cos\left(\phi\right)$	) Coma, $9^{th}$ order
35	9	1	$\left(126R^9 - 280R^7 + 210R^5 - 60R^3 + 5R\right)\sin(\phi)$	) Coma, $9^{th}$ order
36	10	0	$252R^{10} - 630R^8 + 560R^6 - 210R^4 +$	Spherical, 9 <sup>th</sup> order
			$30R^2 - 1$	
37	12	0	$924R^{12} - 2772R^{10} + 3150R^8 - 1680R^6 +$	spherical, 11 <sup>th</sup> order
			$420R^4 - 42R^2 + 1$	

## 8.29.4 Extended Fringe Zernike Polynomial Terms (ZFE)

The extended Fringe Zernike coefficients 1 - 36 are identical to the Fringe Zernike coefficients and have the same order (see table 8.34), so they are not repeated here. The  $49^{th}$  term of the **extended** Fringe coefficients is identical to the  $37^{th}$  term of the Fringe coefficients.

Term	n	m	Extended FRINGE-Zernike-Polynomial	Meaning
37	6	6	$R^6 cos(6\phi)$	Hexafoil, primary X
38	6	6	$R^6sin(6\phi)$	Hexafoil, primary Y
39	7	5	$R^{5}(7R^{2}-6)cos(5\phi)$	Pentafoil, secondary X
40	7	5	$R^{5}(7R^{2}-6)cos(5\phi)$	Pentafoil, secondary Y
41	8	4	$R^4(28R^4 - 42R^2 + 15)cos(4\phi)$	Tetrafoil, tertiary X
42	8	4	$R^4(28R^4 - 42R^2 + 15)sin(4\phi)$	Tetrafoil, tertiary Y
				continued on next page

Table 8.35: Extended Fringe Zernike Polynomials (ZFE)

continued from previous page				
43	9	3	$R^{3}(84R^{6} - 168R^{4} + 105R^{2} - 20)\cos(3\phi)$	Tetrafoil, quaternary X
44	9	3	$R^{3}(84R^{6} - 168R^{4} + 105R^{2} - 20)sin(3\phi)$	Tetrafoil, quaternary Y
45	10	2	$R^{2}(210R^{8} - 504R^{6} + 420R^{4} - 140R^{2} +$	Astigmatism, quinterary,
			$(15)cos(2\phi)$	0 or 90 deg.
46	10	2	$R^{2}(210R^{8} - 504R^{6} + 420R^{4} - 140R^{2} +$	Astigmatism, quinterary,
			$15)sin(2\phi)$	$\pm$ 45 deg.
47	11	2	$R(462R^{10} - 1260R^8 + 1260R^6 - 560R^4 +$	Coma, quinterary, X
			$105R^2 - 6)cos(\phi)$	
48	11	2	$R(462R^{10} - 1260R^8 + 1260R^6 - 560R^4 +$	Coma, quinterary, Y
			$105R^2 - 6)sin(\phi)$	
49	12	0	$924R^{12} - 2772R^{10} + 3150R^8 - 1680R^6 +$	Spherical, quinterary
			$420R^4 - 42R^2 + 1$	
50	7	7	$R^7 cos(7\phi)$	Heptafoil, primary X
51	7	7	$R^7 sin(7\phi)$	Heptafoil, primary Y
52	8	6	$R^{6}(8R^{2}-7)cos(6\phi)$	Hexafoil, secondary X
53	8	6	$R^{6}(8R^{2}-7)sin(6\phi)$	Hexafoil, secondary Y
54	9	5	$R^5(36R^4 - 56R^2 + 21)cos(5\phi)$	Pentafoil, tertiary X
55	9	5	$R^5(36R^4 - 56R^2 + 21)sin(5\phi)$	Pentafoil, tertiary Y
56	10	4	$R^{4}(120R^{6} - 252R^{4} + 168R^{2} - 35)cos(4\phi)$	Tetrafoil, quaternary X
57	10	4	$R^4(120R^6 - 252R^4 + 168R^2 - 35)sin(4\phi)$	Tetrafoil, quaternary Y
58	11	3	$R^{3}(330R^{8} - 840R^{6} + 756R^{4} - 280R^{2} +$	Trefoil, quinternary X
			$(35)cos(3\phi)$	
59	11	3	$R^{3}(330R^{8} - 840R^{6} + 756R^{4} - 280R^{2} +$	Trefoil, quinternary Y
			$35)sin(3\phi)$	
60	12	2	$R^2(792R^{10}-2310R^8+2520R^6-1260R^4+$	Astigmatism, senary 0 or
			$280R^2 - 21)cos(2\phi)$	90 deg.
61	12	2	$R^2(792R^{10} - 2310R^8 + 2520R^6 - 1260R^4 +$	Astigmatism, $\pm$ 45 deg.
			$280R^2 - 21)sin(2\phi)$	
62	13	1	$R(1716R^{12} - 5544R^{10} + 6930R^8 - 4200R^6 +$	Coma, senary X
			$1260R^4 - 168R^2 + 7)cos(\phi)$	
63	13	1	$R(1716R^{12} - 5544R^{10} + 6930R^8 - 4200R^6 +$	Coma, senary Y
			$1260R^4 - 168R^2 + 7)sin(\phi)$	
64	14	0	$(-1+2R^2)(1-54R^2+648R^4-2904R^6+$	Spherical, senary
			$5742R^8 - 5148R^{10} + 1716R^{12}$	

## 8.29.5 Standard Zernike Polynomial Terms (ZRN)

The standard Zernike polynomials are defined according to Born and Wolf [4], and are identical with the first 53 Extended Fringe Zernike terms but are arranged in a different order.

Term	Standard-Zernike-Polynomial	Meaning
1	1	Offset
2	$Rcos(\phi)$	X-Tilt
		continued on next page

Table 8.36: Standard Zernike Polynomials after Born and Wolf (ZRN)

continu	ed from previous page	
3	$Rsin(\phi)$	Y-Tilt
4	$R^2 cos(2\phi)$	Astigmatism $3^{rd}$ order, 0 or 90
		deg.
5	$2R^2 - 1$	Defocus
6	$R^2 sin(2\phi)$	Astigmatism $3^{rd}$ order, $\pm 45$ deg.
7	$R^3 cos(3\phi)$	Triangular-X, 5 <sup>th</sup> order
8	$(3R^3 - 2R)cos(\phi)$	X-Coma and tilt, $3^{rd}$ order
9	$(3R^3 - 2R)sin(\phi)$	Y-Coma and tilt, $3^{rd}$ order
10	$R^3 sin(3\phi)$	Triangular-Y, 5 <sup>th</sup> order
11	$R^4 cos(4\phi)$	Quadratic-X, 7 <sup>th</sup> order
12	$(4R^4 - 3R^2)cos(2\phi)$	Astigmatism, 5 <sup>th</sup> order
13	$6R^4 - 6R^2 + 1$	Spherical and focus, $3^{rd}$ order
14	$(4R^4 - 3R^2)sin(2\phi)$	Astigmatism, 5 <sup>th</sup> order
15	$R^4sin(4\phi)$	Quadratic-Y, 7 <sup>th</sup> order
16	$R^5 cos (5\phi)$	5-fold, 9 <sup>th</sup> order
17	$(5R^5 - 4R^3)cos(3\phi)$	Triangular, 7 <sup>th</sup> order
18	$(10R^5 - 12R^3 + 3R)cos(\phi)$	Coma, 5 <sup>th</sup> order
19	$(10R^5 - 12R^3 + 3R)sin(\phi)$	Coma, 5 <sup>th</sup> order
20	$(5R^5 - 4R^3)sin(3\phi)$	Triangular, 7 <sup>th</sup> order
21	$R^5sin(5\phi)$	5-fold, 9 <sup>th</sup> order
22	$R^6 cos(6\phi)$	Hexafoil, primary X
23	$(6R^6 - 5R^4)\cos(4\phi)$	Quadratic, 9 <sup>th</sup> order
24	$(15R^6 - 20R^4 + 6R^2)cos(2\phi)$	Astigmatism, 7 <sup>th</sup> order
25	$20R^6 - 30R^4 + 12R^2 - 1$	Spherical, 5 <sup>th</sup> order
26	$(15R^6 - 20R^4 + 6R^2)sin(2\phi)$	Astigmatism, 7 <sup>th</sup> order
27	$\left(6R^{6}-5R^{4} ight)sin\left(4\phi ight)$	Quadratic, 9 <sup>th</sup> order
28	$R^6sin(6\phi)$	Hexafoil, primary Y
29	$R^7 cos(7\phi)$	Heptafoil, primary X
30	$R^5(7R^2-6)cos(5\phi)$	Pentafoil, secondary X
31	$(21R^7 - 30R^5 + 10R^3)\cos(3\phi)$	Triangular, 9 <sup>th</sup> order
32	$(35R^7 - 60R^5 + 30R^3 - 4R)cos(\phi)$	Coma, 7 <sup>th</sup> order
33	$(35R^7 - 60R^5 + 30R^3 - 4R)sin(\phi)$	Coma, 7 <sup>th</sup> order
34	$(21R^7 - 30R^5 + 10R^3) \sin(3\phi)$	Triangular, 9 <sup>th</sup> order
35	$R^5(7R^2-6)cos(5\phi)$	Pentafoil, secondary Y
36	$R^7 sin(7\phi)$	Heptafoil, primary Y
37	$R^8cos(8\phi)$	Octafoil, primary X
38	$R^{6}(8R^{2}-7)cos(6\phi)$	Hexafoil, secondary X
39	$R^4(28R^4 - 42R^2 + 15)\cos(4\phi)$	Tetrafoil, tertiary X
40	$(56R^8 - 105R^6 + 60R^4 - 10R^2)\cos(2\phi)$	Astigmatism, 9 <sup>th</sup> order, 0 or 90
		deg.
41	$70R^8 - 140R^6 + 90R^4 - 20R^2 + 1$	Spherical, 7 <sup>th</sup> order
42	$\left(56R^8 - 105R^6 + 60R^4 - 10R^2\right)\sin(2\phi)$	Astigmatism, $9^{th}$ order, $\pm 45$
		deg.
43	$R^4(28R^4 - 42R^2 + 15)sin(4\phi)$	Tetrafoil, tertiary Y
44	$R^{0}(8R^{2}-7)sin(6\phi)$	Hexafoil, secondary Y
		continued on next page

continued from previous page				
45	$R^8sin(8\phi)$	Octafoil, primary Y		
46	$R^9cos(9\phi)$	Nonafoil, primary X		
47	$R^{6}(8R^{2}-7)cos(7\phi)$	Heptafoil, secondary X		
48	$\left(36R^9 - 56R^7 + 21R^5\right)\cos(5\phi)$	Pentafoil, tertiary X		
49	$\left(84R^9 - 168R^7 + 105R^5 - 20R^3\right)\cos(3\phi)$	Trefoil, quaternary X		
50	$\left(126R^9 - 280R^7 + 210R^5 - 60R^3 + 5R\right)\cos(\phi)$	Coma, quaternary X		
51	$(126R^9 - 280R^7 + 210R^5 - 60R^3 + 5R) \sin(\phi)$	Coma, quaternary Y		
52	$\left(84R^9 - 168R^7 + 105R^5 - 20R^3\right)\sin(3\phi)$	Trefoil, quaternary Y		
53	$\left(36R^9 - 56R^7 + 21R^5\right) sin(5\phi)$	Pentafoil, tertiary Y		
54	$R^{6}(8R^{2}-7)sin(7\phi)$	Heptafoil, secondary Y		
55	$R^9sin(9\phi)$	Nonafoil, primary Y		
56	$R^{10}cos(10\phi)$	Decafoil, primary X		
57	$(10R^{10} - 9R^8)cos(8\phi)$	Octafoil, secondary X		
58	$(45R^{10} - 72R^8 + 28R^6)cos(6\phi)$	Hexafoil, tertiary X		
59	$(120R^{10} - 252R^8 + 168R^6 - 35R^4)\cos(4\phi)$	Tetrafoil, quaternary X		
60	$(210R^{10} - 504R^8 + 420R^6 - 140R^4 + 15R^2)cos(2\phi)$	Astigmatism, 0 or 90 deg.		
61	$252R^{10} - 630R^8 + 560R^6 - 210R^4 + 30R^2 - 1$	Spherical, quaternary		
62	$(210R^{10} - 504R^8 + 420R^6 - 140R^4 + 15R^2)sin(2\phi)$	Astigmatism, $\pm 45$ deg.		
63	$(120R^{10} - 252R^8 + 168R^6 - 35R^4)sin(4\phi)$	Tetrafoil, quaternary Y		
64	$(45R^{10} - 72R^8 + 28R^6)sin(6\phi)$	Hexafoil, tertiary Y		
65	$(10R^{10} - 9R^8)sin(8\phi)$	Octafoil, secondary Y		
66	$R^{10}sin(10\phi)$	Decafoil, primary Y		

# 8.30 Zernike Phase Surface

The Zernike phase surface adds terms to the nominal wave front aberration of an optical system. It is most useful for the inclusion of measured interferometer data. Zernike phase surfaces must be defined on surfaces with the same medium on both sides of the surface (preferably AIR/AIR interfaces).

The following examples show definition of the Zernike phase surface, assuming surface 4.

#### In the command line :

```
zrn pha s4! define Zernike phase surfaceinr s4 10! Connects Zernike unit circle to physical aperturezrn s4 c5 0.00123! Zernike coefficient c5 at surface s4 is 0.00123zact s4 c5 1! activate/enable coefficient c5 at surface s4
```

#### In the user dialog:

Invoke the Zernike editor from the menu *Edit / Zernike Coefficients* or from the command line by entering "EDI ZRN" (without the quotes). A dialog box will pop up. The dialog is partially shown in Fig. 8.30.

Check the radio button "**phase**" and enter the appropriate coefficients. Do not forget to activate (enable) the coefficients by checking the "On" field for each coefficient.



Figure 8.46: Editing of Zernike phase coefficients.

# 8.31 User-Defined Surface (UDS)

The user-defined surface allows interrupting the internal ray trace algorithms in OpTaliX and take control of the ray trace. Internally, the ray trajectory is computed up to the surface immediately preceding the user surface, calls a user-written subroutine specified for the surface and then completes the ray trace through the remaining surfaces.

The designation of a surface as user-defined is done by entering the UDS command on that surface or setting the surface type (SUT sk U) directly. Coefficients for the user-defined surface, if any, are defined by the UCO command.

indexUser-defined!surface type	
--------------------------------	--

UDS sij sk	Change surface type to user-defined surface on surface(s)
	sij, respectively surface sk. Alternatively, the sur-
	face type can be set to "U" (see SUT command on page
	68). The UDS surface shape is entirely defined by the
	UCO coefficients (see below) and the user-written subrou-
	tine "usersur.f90" contained in a DLL.
UCO sij sk cij	Coefficient for describing user-defined surface (UDS) type
coefficient	on surface(s) sij sk using the user-written subroutine
	usersur.f90. The maximum number of coefficients is
	91.

#### 8.31.1 Creating a User-Defined Subroutine

The user need only program the (continuous) surface function and the surface derivatives in a FOR-TRAN or C subroutine called "usersur.f90" respectively "usersur.c". Note: The subroutine name must be exactly "usersur", no other name is permitted.

OpTaliX provides a sample subroutine in both FORTRAN and C programming languages, which is kept simple in order to demonstrate the programming interfaces. The sample subroutine defines a parabolic surface. It is found in the directories

```
\optalix\usersur\Fortran for FORTRAN
\optalix\usersur\C for C/C++
```

with appropriate subdirectories for Lahey/Fujitsu FORTRAN, Compaq Visual FORTRAN, Intel Fortran Parallel Studio, and Microsoft Visual C compilers. The source code of the usersur subroutine is given for each language and compiler in sections 8.31.3 to 8.31.6.

The usersur subroutine can also, if needed, call other subroutines or read data files. The subroutine usersur is successively called to iteratively compute the intersection point of a ray with a UDS type surface. After computing the intersection point of the ray with the surface, the surface slope at that point is determined. A special variable icalc must be queried in the usersur subroutine depending on whether the intersection point or the surface slope is to be calculated.

The usersur subroutine that you write in FORTRAN or C must have the following parameters:

```
usersur(icalc,isur,curv,sdata,x,y,z,xn,yn,zn,i_err)
where
```

	Calculation mode (input). Indicates whether to calculate
icala	the surface function or the surface slope.
	1 = calculate surface z coordinate at coordinates x,y
	2 = calculate xn,yn,zn direction cosines at x,y,z
isur	Current surface number for which the function is to be
	evaluated. This is an input parameter which may be used
	to distinguish between various algorithms on different
	surfaces. If only one UDS type surface is used, this pa-
	rameter is normally not needed. See also the note below.
curv	Surface vertex curvature (input). This parameter does
	not have to be used in the usersur subroutine, how-
	ever, its value is also used to calculate first and third or-
	der properties of the optical system.
sdata	Data array with 91 elements for passing data between
	OpTaliX and the usersur subroutine. The elements
	of data correspond to the UCO coefficients C1 to C91.
x,y,z	Coordinates at a point along the ray.
xn,yn,zn	Direction cosines of the surface normal at the point
	(x,y,z).
i_err	Error flag. It should be set to 0 if there is no error gener-
	ated and set to 1 otherwise.

Note: Only one usersur subroutine can be linked to OpTaliX at one time. Therefore all UDS type surfaces in the optical system must use the same usersur subroutine. However, it is possible to program more than one UDS surface description with different coefficients in the same usersur subroutine. The parameter isur designates the surface number currently in use for finding the surface intersection or surface slope. The following FORTRAN sample code illustrates this:

```
if(isur .eq. 3) then
   ! add code for surface 3 here
elseif(isur .eq. 7) then
   ! add other code for surface 7
endif
```

With this technique, there is virtually no limit on the number of different user-defined surface types in an optical system.

#### 8.31.2 Languages and Compilers Supported

Both FORTRAN and C programming languages are supported. The following sections describe the specifics for various compilers. Sample subroutines are supplied with OpTaliX in both languages Fortran and C. These sample subroutines are located in the  $\programming$  language and compiler used.

Creating user defined surfaces is described for the following compilers:

- Lahey/Fujitsu FORTRAN,
- Compaq Visual FORTRAN,
- Intel FORTRAN Parallel Studio
- Intel oneAPI Fortran
- Microsoft Visual Studio

All supported compilers are 32 bit and 64 bit versions. 16 bit versions are no longer supported. All compilers must have version numbers equal or higher as listed below:

Lahey Fujitsu	FORTRAN-95, version 5.7 or later
Compaq/Intel	Visual FORTRAN, version 6.6 or later
Intel Parallel Studio	version 11 or higher
Intel oneAPI Fortran	version 18 or higher
Microsoft Visual Studio	2012 or later

#### 8.31.3 Compiling with Lahey/Fujitsu Fortran 90

Source code example of a user defined surface (UDS) in FORTRAN with specific instructions for the Lahey/Fujitsu compiler:

```
subroutine usersur(icalc,isur,curv,sdata,x,y,z,xn,yn,zn,i_err)
Evaluate the function and its derivatives of a user defined surface
Parameters:
icalc = 1 : calculate surface z coordinate at coordinates x,y (input)
       = 2 : calculate xn, yn, zn direction cosines at x, y, z
      : surface number
: curvature
isur
                                                               (input)
curv
                                                               (input)
sdata(91) : Array containing the user-defined parameters
                                                              (input)
            For example, sdata(1) is the value entered with the
             command UCO C1.
x,y,z : Coordinates of the current position of the ray with
            respect to the origin of the surface
                                                              (input)
xn,yn,zn : Derivatives of the surface at coordinates (x,y,z) (output)
          : Error flag (0 = no error, 1 = error)
i err
                                                              (output)
Notes:
____
The example code given below calculates coordinates and derivatives
of a parabolic surface based on the curvature "curv".
The user will typically substitute his own FORTRAN code for a
particular surface.
More than one surface description can be programmed in this subroutine.
Use the "isur" parameter to distinguish between surfaces and
```

!

!

1

!

1

!

Т

Т

!

!

1

I.

1

!

!

1

Т

Т

!

!

```
determine the interpretation of the coefficients stored in "sdata"
I.
!
      dll export usersur
!
                       :: icalc,i_err,isur
      integer
      double precision :: x,y,z,xn,yn,zn,curv,sdata(91)
      double precision :: fnorm
!
      i err = 0
T
      z = 0.5d0 * curv * (x * x + y * y)
                                   ! surface z-value, paraboloid
T
      if(icalc.ge.2) then
                                    ! calculate surface derivatives at x,y,z
         xn = x*curv
         yn = y*curv
         fnorm = dsqrt(xn\starxn + yn\staryn + 1.0d0)
        xn = xn/fnorm
         yn = yn/fnorm
         zn = -1.0d0/fnorm
      endif
!
      return
      end
```

The parameter list in usersur.f90 is fixed and must not be changed by the user. Compilation and creating a *dynamic link library* (DLL) with Lahey/Fujitsu FORTRAN-95 requires version 5.7 onwards. Note that earlier versions of Lahey/Fujitsu FORTRAN do not create compatible DLL's and libraries.

To create a 32-bit Windows DLL using Lahey/Fujitsu LF95, the -dll switch must be used. Example: LF95 usersur.f90 -dll -win -ml LF90

In order to reference a procedure across a DLL interface, the compiler must be informed of the procedure name and told how to 'decorate' the external names in your DLL. The procedure name is defined by the 'dll\_export' statement in 'usersur.f90'. Note that the procedure name 'usersur' in the 'dll\_export' statement is case-sensitive. It must be written in small letters to be recognized by the OpTaliX main program.

#### 8.31.4 Compiling with Intel Fortran 90 and Compaq Visual Fortran

The Intel Fortran compiler (versions  $\leq 8.xx$ ) and the Compaq Visual Fortran compiler do seamlessly coexist. Current versions tested are Compaq 6.6 and Intel 7.1. here is the source code example of a user defined surface (UDS) in FORTRAN with specific directives for the Intel/Compaq Fortran compilers:

```
subroutine usersur_(icalc,isur,curv,sdata,x,y,z,xn,yn,zn,i_err)
I
!----- for Intel Fortran V7.xx -----
1
     Evaluate the function and its derivatives of a user defined surface
1
     Parameters:
T
     icalc = 1 : calculate surface z coordinate at coordinates x, y (input)
= 2 : calculate xn,yn,zn direction cosines at x,y,z
I
     isur
               : surface number
                                                                 (input)
     curv
               : curvature
                                                                 (input)
     sdata(91) : Array containing the special user-defined parameters (input)
                For example, sdata(1) is the value entered with the
                 command UCO C1.
     x,y,z \qquad : Coordinates of the current position of the ray with
                 respect to the origin of the surface
(input)
     xn,yn,zn : Derivatives of the surface at coordinates (x,y,z) (output)
1
     i_err : Error flag (0 = no error, 1 = error)
                                                                 (output)
```

```
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```

```
1
1
     Notes:
1
T.
     The example code given below calculates coordinates and derivatives
     on a parabolic surface based on the curvature "curv".
1
!
     The user will typically substitute his own FORTRAN code for a
particular surface.
!
1
     More than one surface description can be programmed in this subroutine.
     Use the "isur" parameter to distinguish between surfaces and
!
!
     determine the interpretation of the coefficients stored in "sdata"
1
      !DEC$ ATTRIBUTES DLLEXPORT:: usersur_
      !DEC$ ATTRIBUTES ALIAS: 'usersur_':: usersur_  ! forces lower case
!
                      :: icalc,i_err,isur
      integer
      double precision :: x,y,z,xn,yn,zn,curv,sdata(81)
      double precision :: fnorm
!
      i\_err = 0
!
      z = 0.5d0 \times curv \times (x \times x + y \times y) ! surface z-value (paraboloid)
!
                                   ! calculate surface derivatives at x,y,z
      if(icalc.ge.2) then
        xn = x*curv
         yn = y*curv
         fnorm = dsqrt(xn*xn + yn*yn + 1.0d0)
         xn = xn/fnorm
         yn = yn/fnorm
        zn = -1.0d0/fnorm
      endif
!
      return
      end
```

The parameter list in usersur.f90 is fixed and must not be changed by the user.

**Intel compiler:** Compilation and creating a *dynamic link library* (DLL) with Intel FORTRAN requires version 7.1 onwards. The DLL is created on the command line:

ifl usersur.f90 /LD

**Compaq compiler:** Compilation and creating a *dynamic link library* (DLL) with Compaq Visual FORTRAN from the OS-command line is accomplished by:

DF /dll usersur.f90

Both compilers Intel and Compaq FORTRAN require the following meta instructions:

The procedure name is defined by the '!DEC\$ ATTRIBUTES DLLEXPORT:: usersur\_'directive. Lower case is forced by the alias instruction '!DEC\$ ATTRIBUTES ALIAS: 'usersur\_': usersur\_'.

#### 8.31.5 Compiling with Intel FORTRAN Parallel Studio and Intel oneAPI Fortran

This section describes coding of user-defined surfaces for the "Intel Fortran Parallel Studio" (formerly called "Intel Visual Fortran Compiler"), versions 11.xx onwards, or the Intel oneAPI Fortran, version 18.0 or higher. Here is the source code example of a user defined surface (UDS) in Intel Fortran Parallel Studio:

subroutine usersur(icalc,isur,curv,sdata,x,y,z,xn,yn,zn,i\_err)

!

```
!----- for Intel Visual Fortran Composer, > V9.xx ---- and ------
!----- for Intel one API Fortran compiler, > V18.xx -----
     Evaluate the function and its derivatives of a user defined surface
!
     Parameters:
_____
     icalc = 1 : calculate surface z coordinate at coordinates x, y (input)
!
            = 2 : calculate xn, yn, zn direction cosines at x, y, z
            : surface number
     isur
I
                                                                    (input)
     curv
               : curvature
                                                                    (input)
     sdata(91) : Array containing the special user-defined parameters (input)
                  For example, sdata(1) is the value entered with the
                  command UCO C1.
               : Coordinates of the current position of the ray with
I
     x,y,z
                 respect to the origin of the surface
I
                                                                    (input)
     xn,yn,zn : Derivatives of the surface at coordinates (x,y,z) (output)
I
            : Error flag (0 = no error, 1 = error)
     i_err
                                                                    (output)
T
     Notes:
The example code given below calculates coordinates and derivatives
I
     on a parabolic surface based on the curvature "curv".
     The user will typically substitute his own FORTRAN code for a
I
     particular surface.
More than one surface description can be programmed in this subroutine.
1
I
     Use the "isur" parameter to distinguish between surfaces and
     determine the interpretation of the coefficients stored in "sdata"
!
     !DEC$ ATTRIBUTES DLLEXPORT:: USERSUR
!
                      :: icalc, i_err, isur
     integer
     double precision :: x,y,z,xn,yn,zn,curv,sdata(81)
     double precision :: fnorm
I
     i\_err = 0
T
     z = 0.5d0 \times curv \times (x \times x + y \times y) ! surface z-value (paraboloid)
!
     if(icalc.ge.2) then
                                  ! calculate surface derivatives at x,v,z
        xn = x*curv
        yn = y*curv
        fnorm = dsqrt(xn*xn + yn*yn + 1.0d0)
        xn = xn/fnorm
        yn = yn/fnorm
        zn = -1.0d0/fnorm
     endif
!
     return
     end
```

The parameter list in usersur. f90 is fixed and must not be changed by the user.

Compilation and creating a *dynamic link library* (DLL) with Intel Fortran Parallel Studio requires version 13.xx onwards, and for the Intel oneAPI compiler version 18.xx or higher. The DLL is created on the command line:

ifort /dll usersur.f90

The procedure name is defined by the '!DEC\$ ATTRIBUTES DLLEXPORT:: USERSUR' directive.

#### 8.31.6 Compiling with Microsoft Visual Studio 2012 and higher

A program written in C must bridge the conventions on naming of functions, subroutines and arguments between FORTRAN and C. Since OpTaliX is a FORTRAN package, in the example that follows we will modify the C side accordingly.

The FORTRAN call to the subroutine USERSUR will generate a requirement for an external symbol called \_USERSUR\_. For a subroutine written in C the entry point name must be USERSUR\_ (note the absence of the leading underscore, which will be added by the C compiler).

Typically, arguments in FORTRAN are passed by reference. C compilers, on the other hand, pass scalar variables by value, rather than its address. This essentially means that C functions should be set up so as to expect that all visible arguments are being passed by reference, or as "pointers" in the C lingo (hence the "\*" in front of the variable names).

Also note that all C arrays start at 0 whereas FORTRAN arrays typically start at 1. The parameter adjustment --sdata accounts for this fact.

Notes for C++: C++ allows function overloading. Therefore functions are stored differently in the \*.lib files compared to the classical C. Because we are not overloading any functions here, we instruct the C++ compiler that we want to use traditional C. Note the following code excerpts,

```
#ifdef __cplusplus
extern "C" {
#endif
```

before the usersur declaration, and at the end of the source code

```
#ifdef __cplusplus
}
#endif
```

This makes the linker to store functions correctly regardless of the C compiler used. Here is the sample code of usersur.c, respectively usersur.cpp:

```
#include <math.h>
#include <string.h>
#include <windows.h>
#define PI 3.14159265359
/* Subroutine */
#define usersur_ USERSUR
#ifdef __cplusplus
extern "C" {
#endif
int __declspec(dllexport) usersur_(int *icalc, int *isur, double *curv, double *sdata, double *x, double *y,
                                      double *z__, double *xn, double *yn, double *zn, int *i_err__) {
  /* Builtin functions */
  /* uncomment the following line only if not declared in the math.h file */
  /* double sqrt(); */
  /* Local variables */
  double fnorm:
  /*
         Evaluate the function and its derivatives of a user defined surface */
  /*
        Parameters: */
  /*
         ---- */
```

```
/*
         icalc = 1 : calculate surface z coordinate at coordinates x,y (input) */
  /*
                = 2 : calculate xn, yn, zn direction cosines at x, y, z */
               : surface number
  / *
         isur
                                                                           (input) */
  /*
         curv
                                                                           (input) */
                    : curvature
  /*
         sdata(81) : Array containing the special user-defined parameters (input) */
  /*
                     For example, sdata(1) is the value entered with the */
  /*
                     command UCO C1. */
  /*
        x,y,z___ : Coordinates of the current position of the ray with \star/
  /*
                     respect to the origin of the surface
                                                                          (input) */
        xn,yn,zn % \left( {{{x_{1}},{y_{2}}}} \right) : Derivatives of the surface at coordinates (x,y,z) (output) */
  /*
  /*
        i_err__ : Error flag (0 = no error, 1 = error)
                                                                          (output) */
  /*
        Notes: */
  /*
         ----- */
  /*
        The example code given below calculates coordinates and derivatives */
  /*
         of a parabolic surface based on the curvature "curv". \star/
  /*
        The user will typically substitute his own C code for a */
  /*
        particular surface. */
  /*
        More than one surface description can be programmed in this subroutine. */
  /*
        Use the "isur" parameter to distinguish between surfaces and */
  /*
        determine the interpretation of the coefficients stored in "sdata" \star/
  /* Parameter adjustments */
  --sdata;
  /* Function Body */
  *i_err__ = 0;
  *z__ = *curv * .5 * (*x * *x + *y * *y);
  /* surface z-value (paraboloid) */
 if (*icalc >= 2) {
  /* calculate surface derivatives at x,y,z */
   *xn = *x * *curv;
   *yn = *y * *curv;
  fnorm = sqrt(*xn * *xn + *yn * *yn + 1.);
  *xn /= fnorm;
  *yn /= fnorm;
  \star zn = -1. / fnorm;
 return 0;
}
#ifdef ___cplusplus
#endif
```

The parameter list in usersur.cor usersur.cpp is fixed and must not be changed. All entries after the comment line /\* Function Body \*/ may be freely modified by the user.

Microsoft Visual Studio 2012 or later is recommended. The newer versions allow improved processorspecific optimizations. Creating a DLL using Microsoft Visual Studio is accomplished in several steps:

- 1. From Microsoft Visual Studio select File  $\longrightarrow$  New  $\longrightarrow$  Project.
- 2. Select Win32Project
- 3. Give the project name: usersur
- 4. In the Windows Desktop Project window select application type: Dynamic Link Library (.dll)
- 5. Uncheck the "Precompiled Header"

- 6. Uncheck the "Security Development Lifestyle (SDL)" checks
- 7. In the Solution Explorer → usersur → Source Files, find the code usersur.cpp and delete it.
- 8. Right click the Source Files folder, select Add → Existing item, and add the template usersur.cpp source code copied from the OpTaliX-PRO\usersur\C\MS-Visual-Studio\_2015 directory.
- 9. Select *Configuration Manager* and make sure that Platform setting corresponds to the OpTaliX edition used, i.e., x64 for 64 bit version and Win32 for 32 bit version of OpTaliX.
- 10. Compile your code by selecting  $Build \longrightarrow Build usersur$  (or  $Build \longrightarrow Rebuild usersur$ ). When compilaton is successfull, the Output window reports locaton of created libraries.
- 11. Find the files usersur.lib and usersur.dll in the location above and copy them into the OpTaliX installation directory C:\Program Files\OpTaliX-PRO

It is advised to make backup copies of original usersur.lib and usersur.dll files. OpTaliX will not start if the libraries are not valid.

# 8.32 Lens Modules

A lens module is a black box with defined optical parameter on input and output, but hiding all internal properties and structure. Lens modules are usually selected when the detailed optical prescription is not known or only a conceptual layout of an optical system is required. Only first order properties of a lens can be modelled by a lens module. As a minimum parameter, the module focal length (MFL) must be provided.

MOD sk sij	Converts the surface type of two surfaces into a lens module.
	The surfaces must exist. If only one surface is specified, the
	surfaces sk and sk+1 will be converted.
MFL sk	Module focal length. sk is the first surface of the module range.
mod_focal_length	
MRD sk red_ratio	Module reduction ratio. Note that MRD is the negative magni-
	fication of the module. By default $MRD = 0$ .
MCO sk cij	Module coefficients (reserved for future editions)

A lens module behaves as a *perfect lens* only at a single magnification which is defined by MRD. A lens module must always be defined by two consecutive surfaces of surface type "L". These surfaces define the entrance surface and exit surface of the lens module. Entrance and exit surface represent the principal planes of the module. For thick lenses or lens systems, the separation of the principal planes is defined by the thickness assigned to the entrance surface. All module parameters (MFL, MRD) must be specified at the entrance surface.

Lens modules can be applied only to finite conjugates. Infinite conjugates (object or image space) are approximated. For example, a reduction ratio of zero is modelled internally by  $10^{-16}$ . Similarly, infinite magnifications are treated as  $10^{+16}$ .

Example setting up a lens module:



Figure 8.47: Lens module (perfect lens).

ins	s34	! insert two surfaces which shall define the module
sut	s34 L	! make surfaces 3 to 4 module surfaces by setting surface type to "L",
		! alternatively use the MOD s3 command
mfl	s3 100	! module focal length is 100 mm
mrd	s3 1	! module reduction ratio = 1 (module magnification = -1)

# 8.33 Surface Apertures

Apertures on surfaces are used to define and limit the light beam passing through a lens system. Up to 10 basic aperture shapes (rectangular, elliptical, circular and polygon) can be assigned to a surface. Note that surface apertures must not be confused with the system aperture. For a detailed explanation of defining system aperture see sect. 7.3.5 (page 50).

Each basic aperture on an individual surface may be transmitting or obstructing, it can be decentered in X- and Y-direction from the local surface vertex and it can be rotated. Basic apertures may be logically combined by .and. respectively .or. operators. The operator p is used to address the different basic apertures on a given surface.

REX sij pij [OBS HOL EDG .or. .and.] x_height	Rectangular aperture. x_height is the semi- aperture in X-direction. See also notes below.
REY sij pij [OBS HOL EDG .or. .and.] y_height	Rectangular aperture. y_height is the semi- aperture in Y-direction. See also notes below.
ELX sij pij [OBS HOL EDG .or. .and.] x_half_width	Elliptical aperture. x_half_width is the semi- aperture (half width) in X-direction. See also notes below.
	continued on next page

The following commands define apertures at surfaces:

continued from previous page	-
ELY sij pij	
[OBS HOL EDG .or. .and.]	Elliptical aperture. y_half_width is the semi-
y_half_width	aperture (half width) in Y-direction. See also
	notes below.
	Defines circular aperture radius is the semi-
[OBS HOL EDG .or. .and.]	aperture of the circle. See also notes below
radius	
REC si.j sk pi.j	Defines rectangular aperture x height and
[OBS HOL EDG .or. .and.]	v height describe the semi-apertures in X-
x_neight y_neight	direction and Y-direction respectively. If only
	x height is specified a square aperture is as-
	sumed
APT si., j cir/rec/ell/pol	
	Set aperture type, i.e. the form of a surface aper-
	ture. It can be circular, rectangular, elliptical,
	or a <b>pol</b> ygon. This command is synonymous to
	the "CIR", "ELX", "ELY", "REX", "REY" com-
	mands. It was introduced to facilitate aperture
	shape definitions in a zoom/multiconfiguration en-
	vironment.
ADX sij pij x_offset	X-offset of aperture center
ADY sij pij y_offset	Y-offset of aperture center
ARO sij pij rot_angle	
	Rotate designated aperture on surface(s) sij.
	Rotation is performed after ADX, ADY.
	Polygon aperture. Two forms of defining poly-
	gon vertices are possible: The first form defines
	a single polygon vertex on surface(s) s1],
	aperture element(s) p1 j and vertex (coeffi-
	cient) ck. xk_vertex, yk_vertex are the
	polygon vertex coordinates. Example: pig
PLG sij pij ck xk_vertex	s3 p2 c4 12.0 3.0
yk_vertex	The second form reads all polygon vertices
PLG sij pij file data.plg	from a file data.plg. Note that the "file"
	qualifier in the command is obligatory to inter-
	pret the subsequent string as a file name. The
	(and page 522). See also the details d
	(see page 525). See also the detailed description
	tion 8 22 1) and for reading polygon data (sec-
	a file (section 8 33 1 2)
DEL ADE chici i si ilEDC	Delete aperture definition pi i on aur
א חיזת אני צעוצדיין אדי אני אין אין אין אין אין אין אין אין א	face(s) $c_1$ is the alternate form DET ADE
	skisi i EDG deletes edges on the designated
	surfaces
	54114005.

Notes:

• The parameter p may be omitted for the first sub-aperture, i.e. the commands

```
cir s1 p1 30
cir s1 30
```

are identical.

- OBS means this is an obstructing aperture. Rays which hit the surface inside the border of an obstructing aperture element are blocked.
- HOL denotes a hole at the designated aperture, that is, rays inside a hole aperture are not affected by refraction or reflection on that surface, they "pass through" without any interaction. HOL aperture elements are used with sequential *and* non-sequential surfaces (see also sect. 8.33.2).
- EDG means this is the edge of the element following the designated surface. That is, it is only necessary to specify the EDG for the first surface of an element. EDG values specified on the rear surface of an element are ignored. Element edges are shown in the lens layout plots, are used in weight calculation and in lens element drawings. Edges, however, do NOT generate clear apertures. Use the FHY command instead for defining hard limiting (fixed) apertures.
- EDG apertures are deleted by defining a zero value, for example CIR EDG s4 0, or by the command DEL APE sk|si..j EDG.
- The EDG **option** used in REX, REY, ELX, ELY, CIR or REC commands must not be confused with the EDG **command**, which only defines how edges are drawn in the lens layout plot (VIE).
- By default, apertures do not limit or truncate ray beams, except where an obstructing (OBS) property is specified. However, apertures may limit or truncate beams by defining it "fixed" using the FHY command (see section 8.33.3, page 171 below). Then rays hitting a surface outside the aperture bounds will be blocked.

Examples of aperture shapes are shown below to illustrate usage of the commands:





#### 8.33.1 Polygon Apertures

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Polygon aperture elements are constructed from up to 50 vertices and allow almost arbitrary aperture shapes. Polygon vertices are given as (X,Y) data pairs and are referred to the vertex of the optical surface. The entire polygon can be shifted and rotated by the ADX, ADY and ARO commands. Polygon apertures must be closed, i.e. the last vertex must have the same coordinates as the first vertex. Polygon apertures need NOT to be convex and any shape is allowed as indicated in Fig. 8.48. Up to ten polygon apertures are allowed on each surface, however, the total number of polygon apertures in an optical system is limited to 50.

#### 8.33.1.1 Dialog-based editing of polygon apertures

Polygon apertures are edited in the surface spreadsheet editor (invoked by EDI SUR command) in the "special apertures" tab. Set the aperture type in the first column of this tab to "polygon". The appropriate check box in the last column will be activated. Click on this check box and a dialog box as shown in Fig. 8.48 will be displayed.

The shape of the polygon (but not its absolute size) will always be updated as new vertices are entered. The polygon data can be uniformly scaled respectively a new set of polygon data can be imported from a file.

#### 8.33.1.2 Reading polygon apertures from a file

Complex polygon shapes can also be read in from an ASCII file. The data must be stored as (X,Y) data pairs, the file format must conform to the definition of INT-files as given in section 32.11, page 523. The file extension is preferably .plg, however, any other extension is also accepted. Fig. 8.49 shows an example polygon file of a five-pointed star (note that the first two lines in the file are mandatory):

#### 8.33.2 Hole Aperture

On a "hole" aperture element, rays inside the specified hole aperture are passing through unaffected, i.e. they do NOT undergo refraction, reflection or diffraction on that surface. Hole apertures can be applied to both sequential and non-sequential surfaces. Hole apertures cannot be applied to the base aperture on a surface (i.e. aperture pointer p1), use p2 or higher. Here is a concise command sequence for entering hole apertures:

cirs3p25.0hol! Defines a circular hole on surface 3, aperture element 2, with 5mm radius,rexs4p24.0hol! Rectangular hole on surface 4, aperture element 2, X-height is 4mm,reys4p22.0hol! Rectangular hole on surface 4, aperture element 2, Y-height is 2mm,

Surfa	ce 3 Pu	apil 2	
	X	Y	<ul> <li>Number of data points</li> </ul>
1	10.0000	0.0000	12
2	0.0000	10.0000	_
3	-5.0000	5.0000	
4	-2.0000	3.0000	
5	-4.0000	0.0000	
6	-7.0000	4.0000	
7	-10.0000	0.0000	
8	-10.0000	-5.0000	
9	-5.0000	-5.0000	
10	0.0000	-10.0000	
11	0.0000	-3.0000	· ·
12	10.0000	0.0000	Cash ashara data
13			
14			Import from File
15			
16			
17			Cancel OK
18			•

Figure 8.48: Dialog-based editing of polygon apertures.

Note that special apertures (such as obscurations, holes, polygons, etc.) are **only** active if the the fixed height (FHY) attribute has been assigned to the designated surface. A detailed description on "fixed heights" is given in section 8.33.3.

In sequential systems only, hole apertures are ignored for calculation of the principal properties of an optical system, such as focal length, focus position, aperture ratio, etc., and for all ray aiming purposes. This behaviour assumes that sequential models are primarily based on traditional systems where the imaging function is determined by unobscured lenses/mirrors, and hole apertures were added for modeling additional features. Thus, for determination of system parameters (EFL, BFL, etc.) holes are ignored, whereas in all analysis options holes are correctly taken into account.

In order to study the effects of hole apertures, a simple example has been prepared. Load (restore) the file *\$i\examples\Complex\_Aperture\hole.otx* from the examples directory. A single lens is shown (see Fig. 8.50) bearing two hole apertures on surfaces 2 and 3.

#### 8.33.3 Fixed Apertures (Heights)

It is sometimes necessary to set the aperture radius on a surface to a fixed value which must not change. In a pictorial way, one may say the aperture is "frozen" to a certain dimension. This can be accomplished by the FHY command. Surfaces with fixed apertures are marked by a  $\star$  (asterix) right to the APE-Y column in the prescription listing (LIS command) and in the surface editor. Rays outside the surface aperture marked by FHY are blocked.

Command: plg s3 p2 file c:\star.plg



Contents of file star.plg:

```
Five pointed star

SSZ 1.0 ! scaling factor

11 ! number of polygon vertices

0 1

-0.2245 0.309

-0.9511 0.309

-0.3633 -0.118

-0.5878 -0.809

0 -0.382

0.5878 -0.809

0.3633 -0.118

0.9511 0.309

0.2245 0.309

0 1
```

Figure 8.49: Defining and assigning a five-pointed star polygon aperture from file star.plg to surface 3, pupil number 2.

	Sets the apertures of surfaces si i to fixed
	or floating. Surfaces marked by $FHY = 1$
	block all rays which exceed the aperture ra-
FHY [sij] 0/1	dius. Also, aperture values of these sur-
	faces will not be altered by the program, e.g.
	in modules which automatically set apertures
	(see SET MHT command).
	Automatically determines the maximum re-
	quired surface apertures within the surface
	range sij. The program takes the aper-
	tures of the stop surface and all surfaces
	marked FHY and computes the light beams
	going through the system. All apertures not
	marked FHY will be changed in according to
SET MHT [sij, fij, zij,	the light beam. Note: Ray failures may be re-
over_x, over_v]	ported during maximum aperture determina-
,	tion, for example if total internal reflection oc-
	curs during ray iteration. This, however, will
	be resolved if there is a feasible solution.
	over_x and over_y are the oversizing fac-
	tors for surface apertures (only for lens layout
	plot).
1	

#### **Example:**

Light beams entering the system in Fig. 8.51 are defined by the stop surface (no. 5) and the surface apertures (heights) of surfaces 2 and 7. This way all off-axis beams get vignetted.



Figure 8.50: Hole apertures. Rays inside the hole aperture pass through unaffected. Here shown on a sequential model.

#### 8.33.4 Editing Fixed Apertures in the Surface Editor

The fixed height (FHY) property may be edited in the surface editor in the column right to the APE-Y (aperture height) column:

A fixed (frozen) aperture height is defined by 1 in the \*-column right to APE-Y (corresponds to command FHY sk 1).

Floating apertures are defined by 0 in the \*-column right to APE-Y (corresponds to command FHY sk 0).

# 8.34 Surface Comments

A comment field is provided for each surface, which accepts up to 80 characters of user text. This field is used for improving the readability of the lens data and has no impact on the lens analysis. Surface comments are entered using the command token "COM". For example:

COM s3..4 this is my comment COM s1..2 "this is my comment"

Surface comments are listed by the command LIS COM or together with LIS ALL.

# 8.35 Insert, Invert, Copy, Move and Delete Surfaces



Figure 8.51: Defining vignetting characteristics with fixed apertures.

INS sij target_surf [file file_spec]	<pre>Insert surfaces sij before target surface. The optional pa- rameter [file file_spec] inserts surfaces from a file. Ex- amples: ins s34 ins s34 1 file c:/temp/mylens.otx The second example inserts surfaces 3 to 4 from the file c:/temp/mylens.otx before surface 1 of the current sys- tem.</pre>
INS MIR sk	Insert mirror surface before surface sk. By convention, the sign of radii, thicknesses and aspheric co- efficients are reversed on surfaces following a mirror surface, which can be tedious if done manually. This command auto- matically inserts a surface, converts it to a mirror and reverts all necessary signs on subsequent surfaces. Example: ins mir s3
COP sij target_surf	
[file file_spec]	Copies surfaces si.j to target surface. The target surfaces must exist. The optional parameter [file_file_spec] copies the surfaces from a file. By default, the current directory is searched. Specify the full path if the file resides in a different directory. Examples: copy s34 8! copy surfaces 3-4 to surface 8
[file file_spec]	Copies surfaces si.j to target surface. The target surfaces must exist. The optional parameter [file file_spec] copies the surfaces from a file. By default, the current directory is searched. Specify the full path if the file resides in a different directory. Examples: copy s34 8 ! copy surfaces 3-4 to surface 8 copy s34 8 file mylens.otx ! copy surfaces 34 from file mylens.otx to surface 8 and the following.
[file file_spec]	Copies surfaces si.j to target surface. The target surfaces must exist. The optional parameter [file file_spec] copies the surfaces from a file. By default, the current directory is searched. Specify the full path if the file resides in a different directory. Examples: copy s34 8 ! copy surfaces 3-4 to surface 8 copy s34 8 file mylens.otx ! copy surfaces 34 from file mylens.otx to surface 8 and the following. copy s34 8 file c:\temp\mylens.otx ! As above but surfaces are copied from a file in a directory other than the current directory. The full path must be specified.
[file file_spec] MOV sij target_surf	Copies surfaces si.j to target surface. The target surfaces must exist. The optional parameter [file file_spec] copies the surfaces from a file. By default, the current directory is searched. Specify the full path if the file resides in a different directory. Examples: copy s34 & ! copy surfaces 3-4 to surface 8 copy s34 & file mylens.otx ! copy surfaces 34 from file mylens.otx to surface 8 and the following. copy s34 & file c:\temp\mylens.otx ! As above but surfaces are copied from a file in a directory other than the current directory. The full path must be specified. Move surfaces sij to the position of surface target_surf.

continued from previous page	
DEL sij	Deletes surfaces sij
	Delete mirror surface sk.
	This command combines two operations: It deletes the desig-
DEL MID ch	nated surface sk and reverts all necessary signs on subsequent
DEL MIR SK	surfaces. Surface sk must be a mirror surface, otherwise the
	command is ignored.
	Example: del mir s3
INV sij	Invert surfaces sij

## 8.36 Coatings / Multilayer Stacks

A complete package for design, analysis and optimization of thin film coatings is implemented in OpTaliX. This section describes how predefined coatings may be assigned (i.e. attached) to optical surfaces.

### 8.36.1 Attach Coatings to Surfaces

In the **command line**, attaching coating definitions to optical interfaces (surfaces) is accomplished by the following commands:

ATT sij [ FILE	Attach a multilayer coating to surfaces sij The						
coating_name ]	coating_name refers to a file containing the coat-						
	ing prescription. It must exist. If the option [FILE						
	coating_name] is absent, the default coating (if loaded)						
	will be attached.						
COO sij aut nor inv							
	Orientation of coating when attached to an						
	optical surface.						
	aut = the orientation of the coating stack is						
	automatically determined.						
	nor = normal orientation, i.e. as defined in						
	the coating file,						
	inv = the coating is inverted (for example on						
	a glass-air interface).						
	Example:						
	coo s13 aut						
DEL COA sij	Delete multilayer coating from surfaces sij						

In the **surface editor**, coatings (or multilayer stacks) may easily attached to surfaces by entering the coating file name into the "coating" column of the surface editor, as shown in Fig. 8.53. The corresponding coating file must exist, either in the current directory (i.e. where the current optical design is stored) or in the general coating directory as defined in the program preferences (page 23).

										/	Ape FHነ	rture fixed (frozen) / 1
📢 Su	rface Edi	tor: O:\optalix\s	yste	ms\ACR TES	5T.OTX							
Stand	lard Data	Decenter, Tilts .	Asph	ere GRIN	Solves	Special Aperture	s	Hologram	Mis	c. Array		
	TYPE	Radius		Distance		GLASS		APE-Y	×	Shape		
OBJ	S	0.000000	0	0.1000000E+	-21			0.00	0 0	eircular	ΤI	Aperture free (floating)
STO	S	131.15965	6 v	5.0000	)00	BK7		15.0	1	circular		FHY 0
2	S	-150.80175	0 v	1.5315	507			14.94	4 0	circular 🦯		
3	S	-134.00913	7 v	3.0000	000	SF6		14.80	1	circular		
4	S	-254.13400	6 v	214.10	)43			14.8	0	circular		
IMG	S	0.000000	0	-0.3305800E	-01 v			5.26	50	circular		
EFL = MAG	220.0000 = 0.00000	0 BFL = 21- 0 SYL = 9.5	4.137 53150	3 EPD 17 OAL	) = 30.0 . = 223.	05388 🔽 .6358 🗖	PIN AF	4 0				
Pos.	1 💌	Insert Surf. Ins	ert Fi	e Delete Su	urf.	Help Clo	se					

Figure 8.52: Defining fixed (frozen) apertures in the surface editor.

### 8.36.2 Coating Orientation

Coatings are attached to surfaces as defined in the corresponding coating file. The regular orientation of coatings in OpTaliX is **air - layers - substrate**, respectively for cemented surfaces, **cement - layers - substrate**.

When attaching coatings to specific surfaces, OpTaliX automatically detects the correct orientation of coatings. For example, on an air-glass interface, the coating is attached in normal orientation, i.e. as stored in the coating file, on glass-air interfaces, the coating is automatically inverted. This does not require any user interaction.

In special cases, however, it is advisable to explicitly specify the coating orientation to avoid any ambiguities. For example, cemented surfaces are a good example of overriding the automatic determination. Use the "COO NOR" or "COO INV" commands (without the double quotes), depending on how the layer sequence is defined in the coating file.

A detailed description on creating, changing and optimizing coatings is given in chapter 20 on page 387.

## 8.37 Image Surface Definition

The image surface is typically the last surface in an optical system, however, it can be freely defined by use of the IMG command:

IMG sk

Defines the image surface number. sk must be less or equal the total number of surfaces in the optical system. The IMG command does not change the total number of surfaces in a system. Surfaces greater than IMG are '*inactive*' surfaces (i.e. not included in the ray trace) but are always stored/restored, irrespectively of the IMG setting.

Defining the image surface number is particularly useful in systems with intermediate images. The IMG command allows the re-definition of the image surface and the subsequent analysis and optimization at the new surface with a single command.

Note that the IMG command does not alter the total number of surfaces. That is, moving the image surface to a lower surface number still keeps surface data of **all** surfaces higher than IMG in memory. Also on storing/restoring optical systems, the total number of surfaces in a system is retained, irrespectively of the IMG setting.

For example, the system shown in Fig. 8.54 exhibits an intermediate image. Both the intermediate

(( <sup>st</sup> Su	rface Edi	tor: C:\Temp\	Act	romat.otx											_	
Stand	lard Data	Decenter, Tilts	A	sphere GRIN	So	ves Speci	ial A	pertures H	olo	gram Mis	c.   A	Array				
	TYPE	Radius		Distance		GLASS		APE-Y	×	Shape	GIb	THR	Comment	Coa	ting	
OBJ	S	0.00000000		0.1000000E+21				0.00	0	circular	0	0.00000				
STO	S	131.159656	۷	5.000000		BK7		15.03	0	circular	0	0.00000		AR_1_TE	ST	
2	S	-150.801750	۷	134.2524				14.94	0	circular	0	0.00000		AR_4		
IMG	S	0.00000000		-0.3305800E-01	۷			5.26	0	circular	0	0.00000		4		
<u> </u>																<u>}</u>
EFL =	136.0570	BFL = "	134.	2854 EP	D =	30.05388		🔽 PIM								
MAG = 0.000000 SYL = 5.000000 OAL = 139.2524 C AFO																
Pos. 1 V Insert Surf. Insert File Delete Surf. Help Close																
1			_		_											

Coating name (without extension .otc). Seached first in current directory, then in coating directory as defined in program preferences.

Figure 8.53: Enter coating name on optical surfaces. The coating name corresponds to the coating file name (without the extension .otc). The coating (file) is first searched in the current directory (i.e. where the current optical system resides) and, if not found, in the coating definition directory as defined in the program preferences (page 23).

image and the final image can be simultaneously analyzed/optimized by defining the image surface number separately for each zoom position.

In the surface editor, surfaces greater than IMG are marked by blue colour to indicate that these surfaces are currently not active. Fig. 8.55 gives an example. Notice that parameters of inactive surfaces can always be edited.

There are a few restrictions connected with the IMG command:

- The IMG surface number must be less or equal the total number of surfaces in the optical system.
- The IMG surface number must not be the first surface or the object surface.
- The IMG surface number must always be greater than the stop surface number. If required, move the stop surface to a surface number lower than IMG (for example by zooming the stop surface).



Figure 8.54: Re-defining the image surface number (IMG command) in a zoom/multi-configuration system. Top: Image surface is defined at an intermediate surface (IMG s15). Bottom: Image surface is the last surface in the system (IMG si). The corresponding zoom definitions are shown in the lower right corner (dialog box). The example file is found at:  $i \leq 1 \leq 1$ .



Figure 8.55: Inactive surfaces (i.e. surface numbers greater than IMG sk) are marked by blue colour in the surface editor, but still can be edited.

# Listings, Reports

The LIS command gives an output of a complete lens description of the optical system. The listing also includes the first order properties as obtained from the FIR command.

## 9.1 List Prescription Data

Listings of prescription data and reports are obtained by the command:

LIS [si..j] [ri..j] [options]
or:
LIS [options] > prn|filespec

where options can be one of the following parameter

RAY | GLA | ALG | IND | PIK | CNF | TXT | MUL | OPT | APE | TOL | TPL | COM | CAM | OSP | PAR | DNDT | EXC | ALL

#### Description of list options:

ALL	all options, list everything
ALG	alternative glasses with respect to a base glass. See also sect. 12.5 below.
APE	surface apertures (heights)
CAM	cam parameter.
COM	surface comment
CNF	configuration data
DNDT	absolute dn/dT of selected glasses. See also the notes below.
EXC	Linear expansion coefficient of selected glasses.
	continued on next page

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continued from	continued from previous page					
GLA	Lists all glasses in glass catalogue, which match a specified string. For example, gla bk* = all glasses beginning with "bk" GLA sch:bk* = all glasses from SCHott beginning with "bk" GLA sch:* = all glasses from Schott					
	For example, the pattern $sf*$ lists all glasses beginning with "sf", hence it					
	will list SF1, SF2, SF11, SF6 and so on. The pattern "sf" without asterisk will					
	search for the glass si, which does not exist.					
IND	refractive indices used in current system					
MUL	multilayer definition					
OPT	optimization data					
OSP	optical spectrum					
PAR	paraxial system data. See also FIR (page 250).					
PIK	surface pickups (see also PKL surface pickups)					
RAY	all rays					
REM	remarks					
TOL	tolerances					
TPL	test plate list					

#### Notes:

- The redirection symbol ">" allows immediate text-output to the printer (prn) or graphics output to the printer/plotter (plt) or to a file (filespec).
   Note: The output unit redirection is active only for one single command. Subsequent outputs will then appear on the default output device (screen) again.
- 2. The LIS DNDT command accepts an additional parameter, the temperature (in °C) at which dn/dT shall be calculated. For example, dn/dT data of Schott BK7 glass at 50°C are listed by:

lis dndt bk7 50

Omission of the temperature parameter resorts to the default temperature 20°C. dn/dT data is always listed for wavelengths defined in the system configuration. Glasses or wavelengths where dn/dT data is unavailable return -999.

#### **Command Examples:**

lis	all	! List all relevant surface data
lis	> prn	! Surface listing is redirected to printer (prn)
lis	s15	! List surfaces 1 to 5
lis	ra	! List all rays
lis	r15	! List rays 1 to 5
lis	gla sf*	! List all glasses beginning with "sf"
lis	dndt bk* 50	! List absolute dn/dT for all glasses beginning with "bk" at $50^\circ C$

## 9.2 List Alternative Glasses

Lists alternative (replacement) glasses with respect to a base glass. Alternative glasses are glasses having similar properties on refractive index and dispersion compared to the base glass and therefore may be used to replace the base glass in an optical system. The choice of alternative glasses is based on the given index difference ( $\Delta n_d$ ) and the dispersion difference ( $\Delta \nu_d$ ) at the d-line.

The syntax for listing alternative (replacement) glasses is:

LIS ALG base_glass	List alternative (replacement) glasses with respect to a
[delta_n delta_V] <sup>1</sup>	base_glass. By default, the tolerances on selecting an al-
	ternative glass are $\Delta n_d = 0.001$ on refractive index and
	$\Delta \nu_d = 0.8\%$ on dispersion, however, they may be overwrit-
	ten by specifying delta_n and delta_V. See also the direct
	command 'ALG' (page 201).

Notice that the choice of alternative glasses is solely based on the  $\Delta n_d$  and  $\Delta \nu_d$  differences. It is the designers responsibility to take other glass properties into account, such as partial dispersion, TCE, dn/dT, etc, depending on a particular application. This list is only intended to support you in selecting glasses from alternate vendors.

#### **Example:**

LIS ALG N-BK7

produces the following output:

```
ALTERNATIVE GLASS LIST :
  se glass n_d V_d P(g,F) P(C,s)
SCH:N-BK7 1.516798 64.141 0.5350 0.5612
Base glass
                                        P(C,s)
                                                   TCE
                                                         dndT Melt Price
                                                   7.10
                                                         1.160
                                                               1 1.00
Alternative glasses:
  SCO:BK7 1.516798
                                                                   0.00
                         64.141 0.5350 0.5612
                                                  7.10 1.160
                                                                0
  SCO:UBK7
                1.516800
                         64.264
                                  0.5349
                                         0.5603
                                                   7.00
                                                         1.102
                                                                0
                                                                    0.00
  OHA:S-BSL7
                                 0.5353 0.5601
                1.516328
                         64.116
                                                   7.20
                                                        0.000
                                                                1
                                                                    1.00
               1.516328 64.039 0.5334 0.5646
  OHA:L-BSL7
                                                  5.80 0.000
                                                               0 0.00
  OHA:BSL7Y
               1.516329 64.218 0.5343 0.5636
                                                 6.80 0.000
                                                               1 0.00
  COR:B1664
               1.516802
                         64.198 0.5352 0.5609
                                                 6.80 0.000
                                                               0 0.00
                         64.022 0.5346 0.5594
64.083 0.5358 0.5594
                                                                0 0.00
0 0.00
  SUM:SU-BK7
                1.516328
                                                  0.90
                                                        0.000
  HIK:H-E-BK7
                                                  9.20 0.000
                1.516798
  HOY:BSC7
               1.516797 64.172 0.5343 0.5615
                                                  7.50
                                                       0.541 1 0.00
  CDG:H-K9L
               1.516797 64.172 0.5343 0.5615
                                                 7.50
                                                       0.000 0 0.00
Tolerance on nd
                 : 0.001
Tolerance on Vd
                 : 0.8 %
```

```
Notes:
```

- dndT values are always given as  $10^{-6}$  units
- Melt indicates the glass manufacturers melt frequency. 1 corresponds to very high melt frequency, 5 corresponds to very low melt frequency. 0 means that there is no information available or that the glass is discontinued.
- Price is given relative to SCHOTT BK7. In absence of information, the relative price is 0.00.

<sup>&</sup>lt;sup>1</sup>Note that the previous command 'LIS ALT' is obsolete, however, still supported for backwards compatibility.

## 9.3 Description of Standard Listing Output

The data output with the LIS command are formatted to a fixed number of significant digits. If this is insufficient for a given item of data, full precision can be obtained with the EVA command (see also page 464). There are many options to the LIS command as described in section 9.1, however, the simplest form is just LIS. There are no qualifiers or data associated with the command (except for LIS DNDT, see page 180). You may also wish to direct output to a file with the OUT command (see page 451) prior to applying the LIS command.

The individual data listed with the LIS command, can be listed separately, as described in section 9.1. A standard listing is invoked by the command LIS, which is divided into three parts,

- 1. System data,
- 2. Surface data (standard),
- 3. Paraxial (first order) data.

An example listing (Double-Gauss lens from the examples library) indicates the three-parts logic as shown below:

#### Part 1, System Data:

```
FILE = DOUBLE GAUSS.OTX
                                                                                                  11.Jul.2004
                                                                                                                        15:49
Remarks:
   DOUBLE GAUSS - U.S. PATENT 2,532,751
Wavelength : 0.65630
Weight : 1
                                           0.58760
                                                              0.48610
                                               1
                           1
                                                                         1
REF = 2

        XAN
        0.00000
        0.00000
        0.00000

        YAN
        0.00000
        10.00000
        14.00000

        FWGT
        100
        100
        100

FACT
                       1
                                            1
                                                                     1
PIM = yes
SYM = yes
EPD = 25.0000
```

#### Part 2, Standard Surface Data:

#	TYPE	RADIUS	DISTANCE	GLASS	INDEX	APE-Y	AP	CP	DP	ΤP	MP	GLB
OBJ	S	Infinity	0.10000E+21		1.000000	0.00	С	0	0	0	0	0
1:	>S	28.7249	4.37333	BSM24	1.617644	15.00*	С	0	0	0	0	0
2	S	94.2300	0.14909		1.000000	14.60	С	0	0	0	0	0
3	S	17.4436	6.21211	SK1	1.610248	12.71	С	0	0	0	0	0
4	S	Infinity	1.88848	F15	1.605648	12.26	С	0	0	0	0	0
5	S	10.7346	7.55393		1.000000	8.48	С	0	0	0	0	0
STO	S	Infinity	6.46060		1.000000	7.74	С	0	0	0	0	0
7	S	-13.5175	1.88848	F15	1.605648	8.44	С	0	0	0	0	0
8	S	Infinity	5.41696	SK16	1.620408	10.45	С	0	0	0	0	0
9	S	-17.4934	0.14909		1.000000	11.06	С	0	0	0	0	0
10	S	293.3702	3.42909	SK16	1.620408	11.94	С	0	0	0	0	0
11	S	-31.5576	31.52335		1.000000	12.00*	С	0	0	0	0	0
IMG	S	Infinity			1.000000	12.62	С	0	0	0	0	0

Part 3, Paraxial Data:

PARAXIA	AL DATA AT INFINITE	CONJUGATES:			
EFL		50.00024	SH1	(Princ.Plane 1)	34.36081
FNO		2.00001	SH2	(Princ.Plane 2)	-18.43131
PARAXIA	AL DATA AT USED CON	IJUGATE:			
MAG	(Magnification)	0.00000	SEP	(Entr.Pup.Loc.)	27.93312
NAO	(Num.ape.object)	0.00000	EPD	(Entr.Pup.Dia.)	25.00000
NA	(Num.ape.image)	0.25000	APD	(Exit Pup.Dia.)	28.68792
BFL		31.56893	SAP	(Exit Pup.Loc.)	-25.80720
DEF	(Defocus)	-0.04558	PRD	pupil relay dist	-16.21914
IMD	(Image distance)	31.52335	OAL	(S1->Image)	69.04452
OID	(Object->Image)	0.10000E+21	SYL	(System Length)	37.52117

## 9.4 List Global Coordinates and Global Matrices

Normally an optical system is described with respect to a chain of local coordinate systems for each surface (sequential model). However, it may be desirable to obtain the coordinates of each surface vertex in a global coordinate system. The following commands output the coordinates of surface vertices and the corresponding transformation matrices referred to a given surface.

For reference, see also the related commands for entering surface data referred to another surface (GLO command, page 118).

GSC [sij]	Reports global surface coordinates referred to a reference sur- face which is defined by the GLO command (see below).
GSM [sij]	Reports global surface matrix, referred to a reference surface which is defined by the GLO command (see below). The global surface matrix is a 3 by 4 matrix describing the global tilts and offsets of the surface vertices.
GLO sk [yes no]	Set global coordinates analysis on/off. X/Y/Z surface coordi- nates for SIN, RSI and GSC (see above) are expressed relative to the single global origin defined by GLO. If GLO is not de- fined, sk defaults to s1. If sk is specified, the global surface coordinate output is referred to surface sk, otherwise s1 is used. Examples: glo s3 ! global surface coordinates are referred to surface 3 glo y ! Sets global surface output on. Reference surface is 1. glo yes ! As above, sets global surface output on. Reference surface is 1. glo ! Restore previous sk. If no previous GLO, uses s1. glo no ! Turn off global coordinate output.

Global coordinates of surface vertices may also retrieved from the lens database in EVA commands (page 26.9), in macros (page 457) and in optimization constraints (page 19.7):

XSC, YSC, ZSC	- global vertex coordinates, referred to surface defined by GLO sk.
XSG, YSG, ZSG	- global vertex coordinates, always referred to global system (no surface reference).
CXG, CYG, CZG	- global direction cosines of surface normal

#### Example Output: Global Surface Coordinates (GSC)

Command: gsc

****	***** ABSO	LUTE VERTEX	COORDINATES	RE	EFERRED TO SUI	RFACE 1 **	* * * * * * * * * *
	Surface	vertex coo:	rdinates	:	Direction c	osine of sur	face normal
#	Х	Y	Z	:	NX	NY	NZ
					Alpha	Beta	Gamma
1	0.00000	0.00000	0.00000	:	0.000000	0.0392598	0.9992290
					2.25000	0.0000	0.00000
2	0.00000	-116.19792	-1476.43457	:	0.000000	-0.0155134	0.9998797
					-0.88889	0.00000	0.00000
3	0.00000	-308.74461	273.85521	:	-0.0000020	-0.1651447	0.9862693
					-9.50564	0.00012	0.00000

The GSC command outputs X/Y/Z coordinates of each surface vertex referred to an arbitrary surface (see GLO command), the direction cosine of the surface normals and the global  $\alpha, \beta, \gamma$  Euler tilt angles (in the sequence  $\alpha, \beta, \gamma$ .

#### Example Output: Global Surface Matrices (GSM)

#### Command: gsm

GLOBAL SURFACE VERTEX COORDINATES AND TRANSFORMATION MATRICES:

```
Reference surface = 1
```

#	M11	M12	M13	Х	Alpha	Beta	Gamma
	M21	M22	M2 3	Y			
	M31	M32	M33	Z			
1	1.0000000	0.0000000	0.000000	0.00000	2.25000	0.00000	0.00000
	0.000000	0.9992290	0.0392598	0.00000			
	0.000000	-0.0392598	0.9992290	0.000000			
2	1.0000000	0.0000000	0.000000	0.00000	-0.88889	0.00000	0.00000
	0.000000	0.9998797	-0.0155134	116.197921			
	0.0000000	0.0155134	0.9998797	1476.434571			
3	1.0000000	0.0000000	-0.0000020	0.00000	-9.50564	0.00012	0.00000
	-0.000003	0.9862693	-0.1651447	308.744609			
	0.000020	0.1651447	0.9862693	-273.855207			

Surface tilts and decentrations can be conveniently described by a 3 x 4 matrix of the form:

$$\begin{bmatrix} m_{1,1} & m_{1,2} & m_{1,3} & -X \\ m_{2,1} & m_{2,2} & m_{2,3} & -Y \\ m_{3,1} & m_{3,2} & m_{3,3} & -Z \end{bmatrix}$$
(9.1)

The  $m_{i,k}$  coefficients hold the tilts whereas the fourth column contains the X/Y/Z decentrations of the surface vertex with respect to the chosen reference. For a more detailed explanation of tilts defined by matrix notation see also section 8.19, page 115. In addition the  $\alpha, \beta, \gamma$  Euler tilt angles (in the sequence  $\alpha, \beta, \gamma$  are listed in the rightmost three columns.

## 9.5 List User-Defined Variables

LVR	Allows output of information about user-defined variables. Lists the current
	variable names and the associated arguments (numeric values or string).
	See also definition of variables in section 26.11, page 465.

## 9.6 List User-Defined Functions

LFC	Allows output of information about user-defined functions.	Lists the cur-
	rent function names and the associated function definitions.	See also defi-
	nition of functions in section 26.16, page 470.	

# Lens Layout Plot

10

Plots the optical system as a cross-section or 3-D perspective drawing. The command accepts optional parameters to control the type of representation. See also the GRA command (section 25.1, page 452) for output to the printer and for export to other graphics formats.

	Plots cross-section or perspective view of lens layout. sec is a single character describing the type of layout plot (op- tional):
	X : cross section in X/Z plane
	Y : cross section in Y/Z plane
VIE	P : perspective view (wire frame)
[sec sij zk scale ?]	sij = surface range, e.g. s37, (optional)
	zk = zoom position (optional)
	<pre>scale = plot scale (optional)</pre>
	? invokes a dialog box to edit lens plotting parameters.
	Example command: vie Y s37 z4 0.5
VPT azimuth elevation	Defines the azimuth and elevation angles (in degree) for
	three-dimensional perspective plot. The azimuth angle is
	measured in the X/Z-plane from $-180^{\circ}$ to $+ 180^{\circ}$ , with $0^{\circ}$
	directing to the -X axis. The elevation angle is measured
	in the X/Y-plane, ranging from $-180^{\circ}$ to $+180^{\circ}$ . The per-
	spective distance is always at infinity (parallel projection).
	The graphics window containing the perspective plot will be
	automatically updated if it is opened.
LDS	Same as VIE, however, the layout plot is always drawn in
	a screen window, irrespective of other settings of graphics
	output units. See also setting of other graphic output units
	by the GRA command, page 452.
	continued on next page

continued from previous page	
REN	Create an almost photo-realistic rendered image of the lens system. The rendering information is written to the file "optix.pov" in the $OpTaliX$ temporary directory (usually /optix/temp) and the POV rendering engine is subse- quently called. See also section 10.1 on how to interface OpTaliX to POV. The rendering information (POV-file) may also be separately written (exported) to a specific file using the EXP_POV command (see page 499)
RSP	Traces a single ray in the Y/Z lens layout plot. The start coordinates of the ray can be interactively adjusted in field and aperture using slider bars in a dialog box. This command does not output any ray trace data. Use the command RSI on page 240 to obtain precise ray coordinates.
AAP yes no	Plots asymmetric apertures. In lens plot, draws only the used aperture of a surface. AAP no plots the full surface aperture, irrespective of the actual area used by the light beams (surfaces are drawn symmetrical to their local axis). AAP no is the default.
POX,POY,POZ [zij zk]	Plot offsets (in paper coordinates). Shifts the lens layout plot in x- and y-direction on the paper. For "zoomed" systems, individual values for POX,POY,POZ may be specified. In this case, the plot offsets must be preceded by a ZOO qualifier and specified as described in the zoom section (see page 194).
EDI LDR	Edit lens draw parameter for lens layout plot. A dialog box is invoked.
PPOS plot_pos	Plot zoom position. This is an extended variant of the POS command for setting a specific zoom position. If plot_pos, an integer number between 1 and the maximum defined zoom positions, is specified, only the layout of position plot_pos will be drawn. If plot_pos is 0, <i>all</i> positions will be plotted.
	continued on next page

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	Edge d ements number (edge_s of the va	rawing. are drawr (edge_ty string). rious edge t	Specifies how edges of lens el- n. Edges may be specified by rpe_no) or by a descriptive string See also Fig. 10.1 for an explanation types.
	edge	edge	
	type	string	
		yes	Edges are drawn on all elements for
EDG [sij yes no] edge_type_no or EDG [sij yes no]	0	no	which edge_type_no is non-zero, Without surface specifier, omits drawing of <i>all</i> edges, only surfaces are drawn on elements, with surface specifier, omits draw- ing of edges only for the specified
edge_string			surfaces,
	1	lin	connects edges linearly,
	2	ang	connects edges by angled facets (default),
	3	rec	connects edges by rectangular facets.
	Example edg s5	e: 3 or edg	s5 rec ! Draws edges on lens ele-
	ment as 1	rectangular	tacet.

#### **Examples:**

vie	y s15 2.5	Lens draw, Y/Z-section, surfaces 1-5, scale = $2.5$
vie	1.5	Lens draw, scale = 1.5, the other parameters are taken from the pre- vious settings.
vie	0	Plot scaling is automatic. The program internally adjusts the plot scale to fit the layout plot onto the paper.
vie	?	Invokes a dialog box for adjustment of plot parameters prior to layout plotting.
edg	s5 3	Draws edges on lens element as rectangular facet.
edg	s5 rec	As above, draws edges on lens element as rectangular facet.

## **10.1 Using POV Rendering Engine**

Creating photo-realistic pictures is accomplished by invocation of the Persistence of Vision (POV) renderer. POV is free and may be downloaded from http://www.povray.org. It must be installed separately and OpTaliX provides an interface to POV via the export module. In order to tell OpTaliX the location of POV, the path to the rendering engine must be modified in the OpTaliX configuration file optix.cfg. This may be accomplished in two ways:

1. Modify the file optix.cfg, which resides in the OpTaliX installation directory. Search for the key-word RENDER and change the path accordingly. Path names containing blanks must be enclosed in apostrophes. A typical example is



Figure 10.1: Various types of edge drawing.

RENDER = "c:/pov31a/bin/pvengine.exe"

2. From the main menu, select *FILE* -- > *PREFERENCES*. A dialog box appears to modify default search paths. The path to POV may be entered directly into the appropriate field or searched by clicking on the button right to the path-field.

**Information:** In order to use the POV interface, OpTaliX must be installed on a writeable medium. If OpTaliX is executed from a non-writeable medium (a CD\_ROM for example), the whole OpTaliX tree must be copied to a medium, which has write access.

## **10.2** Plot Rays

Only for purposes of plotting the lens layout, a set of special rays (hereafter denoted as *plot rays*) may be generated and stored with the optical system. These rays, however, are completely independent from rays generated internally by the program for image analysis.

Plot rays are generated by the following commands:

SET RAY	Generates a set of standard plot rays. These are typically 5 rays per field point: - a chief ray going through the stop center ( or the entrance pupil center depending on the ray aiming method RAIM), - a meridional (tangential) upper limit ray - a meridional (tangential) lower limit ray - a sagittal upper limit ray - a sagittal lower limit ray.
SET FAN [Y] [num_fan_rays]	Sets a fan of rays in Y-direction. The number of rays (num_fan_rays) is uniformly distributed across the entrance pupil. Vignetted rays are not shown. Omission of the optional parameter Y or num_fan_rays uses the previous setting or the default setting (11 rays across aperture in Y- direction).
	continued on next page

continued from previous page			
SET FAN [X] [num_fan_rays]	Sets a fan of rays in X-direction. The number of rays (num_fan_rays) is uniformly distributed across the entrance pupil. Vignetted rays are not shown. Omission of the optional parameter X or num_fan_rays uses the previous setting or the default setting (11 rays across aperture in Y- direction).		
SET FAN [XY] [num_fan_rays]	Sets a fan of rays in both X-direction and Y- direction. The number of rays (num_fan_rays) is uniformly distributed across the entrance pupil. Vignetted rays are not shown. Omission of the optional parameter XY or num_fan_rays uses the previous setting or the default setting (11 rays across aperture in Y-direction).		
SET FAN [C] [num_circ_rays]	Sets a fan of rays uniformly distributed around the used aperture circumference. Vignetting of the entrance beam is considered, thus, the plot rays may become elliptical in shape. Omission of the optional parameter C or num_fan_rays uses the previous setting or the default setting (11 rays across aperture in Y-direction).		
RAYX rij abs_X_value	Absolute start coordinate X in entrance pupil for plot ray(s) ij.		
RAYY rij abs_Y_value	Absolute start coordinate Y in entrance pupil for plot ray(s) ij.		
RAYCX rij cosine_x	Direction cosine in X-direction in the entrance pupil for plot ray(s) ij.		
RAYCY rij cosine_x	Direction cosine in Y-direction in the entrance pupil for plot ray(s) ij.		
DEL rij	Deletes plot rays ij.		
DEL ra	Deletes all plot rays.		

**Note:** Ray definitions may be overwritten, if automatic ray generation is checked in the lens layout plot (see command EDI LDR).



Figure 10.2: Examples of generating plot rays.

## 11

# **Zoom and Multi-Configuration**

The term "zoom" is used throughout the manual as a generally accepted synonym for "multiconfiguration" systems (bearing in mind that classical zoomed systems mainly alter the air-space between lenses while true multi-configuration systems allow the modification of *any* parameter). Thus, in "true" multi-configuration systems, the lens can be used at different wavelengths, different tilt/scan angles, different object fields, to name a few.

The zoom features are:

- Almost any lens data parameter which can be edited may be zoomed
- all zoom data are saved as part of the lens,
- "dezoom" lens data to any selected zoom position

A zoom or multi-configuration system is set up by the following steps:

- 1. Define the number of configurations
- 2. Define the parameter for each zoom configuration
- 3. define the optimization parameter for each configuration (if any)

Each step is described in detail in the following sections.

#### **11.1** Number of Zoom Positions

The number of zoom positions in OpTaliX is theoretically unlimited, however, there may be practical limitations imposed by your hardware configuration. The number of zoom positions is set by the command

```
ZOO n_pos
```

with  $n_{pos} = number of zoom positions$ .

## **11.2 Define Zoom Parameter**

A "zoomed" parameter always requires a preceding ZOO qualifier, if entered from the command line. For example, to make the thickness at surface 3 variable in a zoom/multiconfigurationn systems, the command would be:

#### ZOO THI S3 1.0 12.0 16.0

The number of parameter must match the number of zoom positions entered by the  $ZOO n_pos$  command. If the number of variables entered is less than the number of zoom positions, then the remaining variables are assumed zero (0).

Also note the command EDI ZOO which invokes a spreadsheet-like editor to define zoom/multi-configuration parameters (sect. 11.3).

The command syntax is:

ZOO n_pos	Define the number of zoom positions.
EDI ZOO	Edit zoom parameter. Invokes a spreadsheet editor.
ZOO operand	Converts a non-zoomed parameter into a zoomed parameter.
parameter_1	"operand" can be any $OpTaliX$ -command, "parameter"
parameter_n	any value appropriate for the operand. Examples are given be-
	low this table.
ZED	Text based editor for editing zoom parameters. This option is <i>only</i> recommended if more than 100 zoom positions or more than 250 zoom parameter rowws/lines shall be handled. Otherwise use the "EDI ZOO" command explained above. The ZED command invokes an ASCII editor for modifying zoom position parameters in a command-like fashion.
POS zoom_pos	Sets a zoomed system to the zoom position "zoom_pos", which is then the current zoom position. All subsequent per- formance analysis (e.g. MTF, PSF, etc) are performed at the currently selected position. It is important to note, that the over- all zoom parameter are not destroyed (as in DEZ command, see below). Example: POS 3 selects the current zoom position 3. A subsequent sys- tem listing (LIS-command) or a MTF-analysis will then be performed at zoom position 3.
	See also the PPOS command on page 188 for plotting only one specific zoom position.
DEZ zoom_pos	Dezoom: Freezes a zoomed system to a non-zoomed (single position) system at the position "zoom_pos". All zoom parameter are lost.
ZOO POX value(z1) value(zn) ZOO POY value(z1) value(zn) ZOO POZ value(z1) value(zn)	Set the plot offset for each zoom-position referred to the center of the paper plotting area. The offset values are given in mm. These commands were introduced to place the lens layout plots (lens drawings) on the paper for each zoom position individu- ally. Example: zoo poy 80 40 0 -40 -80 ! Plots the lens layout plots for the zoom positions 1-5 vertically in Y-direction on the paper, that is position 1 is plotted 80mm above the paper center, position 2 is plotted 40mm above the paper center, and so on.

**Examples:** 

Z00 Z00	3 THI s2 2 4 6	Select 3 zoom positions Zoom thickness s2 is 2mm, 4mm, 6mm at position 1 to 3
ZOO	ADE s36 10 20 30	Zoom X-tilt of surfaces 3-6 to values 10, 20 and 30 degree at positions 1 to 3
DEZ	2	"Dezooms" a system to a non-zoomed system at position 2. For the example given above, the following fixed set- tings are selected: THI s2 4, and ADE s36 20
ZOO	STO s1 s4 s6	Zoom stop surface.
Z00	STO 1 4 6	as above, but without explicit surface qualifier.
ZOO	GLA s1 bk7 sf6 f2	zoom glasses

## 11.3 Spreadsheet Zoom Editor

Zoomed parameter may also be conveniently entered in a spreadsheet like editor. The zoom spreadsheet editor window is capable of displaying and editing up to 50 zoom/multiconfiguration positions. If more than 50 positions are needed, enter zoom parameters in the command line or use the text base zoom editor (ZED command). The zoom editor spreadsheet is invoked by the command

EDI ZOO

Each parameter in the editor is displayed in a separate cell. For example, three fields (YAN) and three axial separations (THI) are zoomed in the examples file

\$i\examples\zoom\laikin-35-1.otx. In the command line, the zoom parameters would be
entered as

```
zoo 4
zoo yan f1 0 0 0 0
zoo yan f2 15.0 7.0 3.0 1.5
zoo yan f3 28.0 14.0 6.5 3.05
zoo thi s5 0.133000E+01 0.2435000E+02 0.4013000E+02 0.5095000E+02
zoo thi s10 0.5688000E+02 0.3234000E+02 0.1431000E+02 0.1000000E+00
zoo thi s15 0.4300000E+00 0.1950000E+01 0.4210000E+01 0.7600000E+01
zoo poy 70 20 -20 -70
```

and in the zoom spreadsheet editor as shown in Fig. 11.1.

Notice that there is a limit on the maximum number of zoom parameter entries (rows/lines) in the spreadsheet zoom editor. Currently only 120 zoom parameter lines are accepted. This limit is only defined to limit system resources and allow OpTaliX to be run also on computers with limited memory.

The first column, labelled "VARIABLE", always holds the parameter to be zoomed. This can be any parameter describing the optical system such as curvatures (CUY), radii (RDY), distances (THI), tilt/decenter (XDE, ADE, ...), wavelength (WL), aperture (EPD,NA,NAO) and so on. Any parameter which can be changed in the command line will also be accepted in the zoom editor.

The second column, labelled "SUR/FLD" specifies surface number or field number or wavelength number. Since the cells in the zoom editor are a direct representation of the (string) parameters entered in the command line, a corresponding surface or field or wavelength letter symbol must preceding.

(Cal Z	oom/Multico	onfiguration	Data			_ [	1 ×
#	1 = 1						
	VARIABLE	SUR/FLD	Pos. 1	Pos. 2	Pos. 3	Pos. 4	-
1	YAN	F1	0	0	0	0	7
2	YAN	F2	15.0	7.0	3.0	1.5	
3	YAN	F3	28.0	14.0	6.5	3.05	1
4	THI	S5	0.1330000E+01	0.2435000E+02	0.4013000E+02	0.5095000E+02	
5	THI	S10	0.5688000E+02	0.3234000E+02	0.1431000E+02	0.1000000E+00	
6	THI	S15	0.4300000E+00	0.1950000E+01	0.4210000E+01	0.7600000E+01	
7	POY		70	20	-20	-70	7-
-	1	1	1	1			-
Row	1	Column	1				-

Figure 11.1: Zoom Editor window, showing the zoom parameters on the example of  $i\geq 1.0$ 

Thus, like in the command line, surface 3 is specified as "s3" (without the quotation marks) in the corresponding cell. Field number 2 would be specified as "f2" and wavelength number 4 as "w4".

All subsequent columns hold the parameter data for each zoom position.

#### Notes:

There are a few parameters which are not dependent on either field, surface or wavelength. These are 'PIM', 'POX', 'POY', 'POZ', 'DEF', 'EPD', 'FNO', 'NA ', 'NAO', 'MAG', 'RED', 'STO', 'WRX', 'WRY', 'ZWX', 'ZWY', 'RCX', 'RCY', 'M2 ', 'MFR'. For these cases the corresponding cell in the second column is greyed, indicating that no entry is required in this cell.

Analysis options such as MTF, PSF, etc) are always calculated at the currently selected zoom/multiconfiguration position. Thus, to do performance analyses for various zoom positions, the corresponding zoom position must be selected prior to the dedicated analysis. The zoom position is set by the command "POS i" where "i" is the zoom position. A few options such as spot diagram (SPO), rim ray fan (FAN) and lens layout (VIE) are designed to plot *all* positions in one graph.

## 11.4 Insert, Copy, Delete Zoom Positions

INS zij	Insert zoom positions zij. Zoom data at higher position numbers will be shifted accordingly.
DEL zij	Delete zoom positions zij. Zoom data at higher position numbers will be shifted accordingly.
COP zk target_pos	Copy zoom position zk to target_pos. This command overwrites data at the new position (target_pos). If re- quired, insert a new zoom position (INS zij) prior to copying zoom position data. Only one position can be copied at a time.

Zoom positions may also be inserted or deleted from the zoom editor window by clicking on the appropriate icons in the zoom editor toolbar as shown in Fig. 11.1. An explanation of the icons is given below.



## **11.5** Text based Zoom Editor

In addition to the spreadsheet zoom editor, a text based editor for zoom/multiconfiguration data is available. This option is offered because the spreadsheet zoom editor is currently limited to 120 parameter definitions (rows/lines). The reason is caused by the fact that the number of cells in a grid editor corresponds to the system resources. The larger the grid, the more system resources are required. In order to allow OpTaliX to be run on computers with limited memory, this limitation has been deliberately defined.

However, the number of zoom/multiconfiguration parameters that can be edited in the *text based* zoom editor is unlimited. The text based zoom editor is invoked by the command

ZED Invoke text based zoom/multiconfiguration editor. A spreadsheet zoom editor, if opened, is automatically closed.

This command opens an editor window similar to figure 11.2.



Figure 11.2: Text based Zoom Editor, showing the zoom parameters on the example of  $i\$  si\examples\zoom\laikin-35-1.otx. See also the command "EDI ZOO" which displays the spreadsheet zoom editor (default).

## 11.6 Solves in Zoom Systems

Solves are active **only** in the first zoom position. The solved parameter is then unchanged for remaining positions.

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## 12

# **Tools and Utilities**

#### 12.1 Autofocus

Finds the best focus of an optical system by adjusting the back focal distance or any other selectable axial separation. It provides an easy and quick means to put the image plane in focus. There are several function types according to which the focus is determined: minimum rms-spot size (also in X- or Y-direction), minimum wavefront error, maximum MTF or maximum coupling efficiency. The best focus location depends upon the criterion selected. Focusing can be accomplished at selected fields and wavelengths or as an average over the full field. For zoom systems, focusing is always performed at the currently selected position (see POS command).

Since only axial separations are altered, autofocus does not account for a tilted image plane. Adjusting the image plane tilt as well (for instance in non-symmetric systems) requires optimization by proper setting of surface tilts ADE, BDE, CDE as variables.

AF function_type [ fij   wij   si   ? ]		
Searches best focus (autofocus) at selected fields and wavelengths by		
adjusting the axial separations (thicknesses). By default, the back focus will		
be adjusted. In case of "PIM yes", the defocus (DEF) is changed. In case		
of "PIM no", autofocus uses the axial separation of the last surface. In case		
a dedicated surface is specified (eq. sk), the axisl distance (thickness) at this		
surface is used to adjust the best focus.		
function_type is one of the 3-character strings:		
CDD spot diameter rms		
SPD spot diameter, mis		
SPX spot diameter, rms, in X-direction only		
PY spot diameter, rms, in Y-direction only		
WAV wavefront error, rms		
MTF modulation transfer function (MTF). The spatial frequency, at.		
which MTF-autofocus is performed, is set by AFR (see page 271),		
or below		
CEF Coupling efficiency.		
AFR autofocus_frequency Spatial frequency used in AF command (see above). It is		
given in Lp/mm for focal systems, in Lp/mrad for afocal		
systems		

#### **Examples :**

af	Autofocus without any parameter adjusts the back focus (default) for all wave- lengths and fields at the currently selected zoom position.
af ?	invokes a dialog box to select from various autofocus options.
af spd f13 w3	determines the best focus for minimum rms-spot diameter at fields 1-3 and wavelength number 3.
af mtf s4 f1	searches best focus on the basis of maximum MTF at field point 1 and uses thickness 4 as variable.
afr freq	Sets spatial frequency for autofocus optimization to freq, in Lp/mm for focal systems, respectively Lp/mrad for afocal systems. This setting does not affect analysis frequencies, such as MFR, MFRD, MFRF.

## 12.2 Scaling

Scales the optical system (or part of it) by a defined factor. The command syntax is

SCA sij scale_factor	Scale range of surfaces sij by scale_factor.
SCA sa scale_factor	Scale entire system (sa = all surfaces) by
	scale_factor.
	Scale entire system by specifying a target value for
	either EFL, OID, SYL, EPD or OAL.
SCA [EFL OID SYL EPD OAL]	Example:
target_value	sca efl 100 ! Scales entire system such that
	a focal length (EFL) of 100mm is obtained.

## 12.3 Invert System

Inverts the optical system (or part of it). Parameters, which describe the usage of the system (aperture, field, etc.), however, are not altered.

INV sij	Invert (reverse) a range of surfaces sij.

## **12.4** Convert fictitious Glasses to real Catalogue Glasses

Converts a fictitious glass to a catalogue glass (a "regular" glass). Fictitious glasses are characterized either by a 6-digit MIL-number as described on page 229 or by DNO or DVO offsets (see page 237). The conversion searches for a nearest glass in the glass catalogues, based on  $n_d$  and  $\nu_d$ . Partial dispersions are not taken into account.

There exist special glasses (like gradient index glasses, "infrared" glasses) for which no valid MIL representation exist. In this case the program will not return meaningful results.

REG [sij   cat_code1	Convert a fictitious glass to a regular cata-
cat_code10   ? ]	logue glass by searching the nearest glass in
	the $n-\nu$ domain (glass map). The cat_code
	is a three character short code identifying the
	manufacturer. The allowed short codes are
	found in table 13.2 (page 224). Up to 10 cata-
	logue codes may be specified simultaneously.
	Examples:
	REG sa SCH : replace all fictitious glasses
	by nearest Schott glasses.
	REG s25 HOY HIK : replace fictitious
	glasses on surfaces 2 to 5 by nearest catalogue
	glasses from Hoya or Hikari.

The catalogues to be searched for a nearest glass may also be conveniently selected in a dialog, accessible from the main menu "Tools" --> "Fictitious glass to catalogue glass" as shown in Fig. 12.1. Select all glass catalogues that apply.

📢 Search for nearest catalogue glass 💶 🗙						
Convert a fictitious glass by searching for the nearest catalogue glass. Select the catalogues below. Multiple selections allowed.						
Schott 2000						
Old Schott						
🔲 Ohara						
🔽 Hoya						
Corning						
🔲 Sumita	Cancel					
🔲 Hikari						
🗖 Chinese	OK					

Figure 12.1: Select glass catalogues for converting fictitious glasses to regular catalogue glasses.

## **12.5** Find Alternative Glasses

Find alternative (replacement) glasses from a different vendor with respect to a base glass. Alternative glasses are glasses having similar properties on refractive index and dispersion compared to the base glass and therefore may be used to replace the base glass in an optical system. The choice of alternative glasses is based on the given index difference ( $\Delta n_d$ ) and the dispersion difference ( $\Delta \nu_d$ ) at the d-line. Hence, alternative glass finding is valid only for the visible (400-700nm) spectral range.

ALG base_glass [delta_n delta_V]	Find alternative (replacement) glasses with respect to a base_glass. By default, the tolerances on selecting an alternative glass are $\Delta n_d = 0.001$ on refractive index and $\Delta \nu_d = 0.8\%$ on dispersion, however, they may be overwritten by specifying delta_n and delta_V.
----------------------------------	----------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------

Notice that the choice of alternative glasses is solely based on the  $\Delta n_d$  and  $\Delta \nu_d$  differences. It is the designers responsibility to take other glass properties into account, such as partial dispersion, TCE, dn/dT, etc, depending on a particular application. This list is only intended to support you in selecting glasses from alternate vendors.

## 12.6 Weight and Volume

This option calculates the weights, volumes and center of gravity of lenses in the optical system. Only the glass weight of the system is included, mechanical spacers and housing are ignored. The volume of spherical lenses with circular base aperture is calculated analytically. Aspheric surfaces and lenses with rectangular or elliptical base aperture are integrated numerically. The weight is computed from the specific gravity of the material as stored in the glass catalogues.

The diameter of the lens is taken from the maximum surface aperture (see sect. 8.33), independent of whether they are checked (fixed aperture) or not. The edge of the surface with the smaller aperture is squared up to the larger aperture.

If edges are specified (see EDG option in section 8.33), they define the enclosed volume. Use of EDG apertures allow the definition of 'edge allowances', or to match values assigned from the housing design.

The weight of front surface mirrors can be calculated provided thickness and specific gravity of the mirror are supplied using the THM and SPG commands (see table below). The back surface of front surface mirrors is always assumed plano.

WEI [sk sij]	Compute weight and volume of lenses. Includes aperture obscurations and holes. Tilted surfaces are not supported. For mirror surfaces, check also the commands THM and SPG for setting mirror thick- ness and specific gravity of mirror material.
SPG [sk sij] gravity	Specific gravity in $g/cm^3$ . This command overwrites any pre-defined value stored in the glass catalogues. Enter SPG sk sij 0 to delete any user-defined specific gravity data.
THM [sk sij]	Center thickness of mirror. This command has no
mirror_thickness	influence on the construction parameter, it is only
	required for weight calculation and for ISO element
	drawing of mirrors.

#### Example 1:

The following example is a standard double Gauss lens, taken from the examples library

\optix\examples\misc\double\_gauss.otx as shown in Fig. 12.2. It also indicates how edges are assumed in the WEI option.



Figure 12.2: Double-Gauss example, showing edges used for weight calculation.

The output table contains surface and element number, volume, specific gravity, weight and center of gravity. The centers of gravity given for the individual lenses refer to the vertex of the front surface, whereas the center of gravity for the entire system is referred to the first surface of the system.

WEIGHT	CALCULATION:						
	Element	Volume	Gravity	Weight	Cente	er of Grav	ity
Surf.	Number	(cm^3)	(g/cm^3)	(g)	Х	Y	Z
1-2	1	2.05929	6.300	12.974	0.000	0.000	3.280
3-4	2	1.84480	3.560	6.567	0.000	0.000	4.052
4-5	3	2.34401	3.480	8.157	0.000	0.000	2.676
7-8	4	1.31742	3.480	4.585	0.000	0.000	-0.163
8-9	5	1.35685	3.580	4.858	0.000	0.000	1.947
10-11	б	0.96652	3.580	3.460	0.000	0.000	1.299
	Total :	9.88889		40.600	0.000	0.000	16.629
Notes:	Center of grav Center of grav	ity of lenses	s are referre system is re	d to the fi ferred to i	ront surface first surfac	e of each	element.

We will now make all surfaces aspheric (use command sut sa a), which forces 2-D numerical integration. Volume and weights of the elements are slightly different due to the numerical integration.

	Element	Volume	Gravity	Weight	Cente	er of Grav	ity
Surf.	Number	(cm^3)	(g/cm^3)	(g)	Х	Y	Z
1-2	1	2.05960	6.300	12.975	0.000	0.000	3.280
3-4	2	1.84512	3.560	6.569	0.000	0.000	4.052
4-5	3	2.34416	3.480	8.158	0.000	0.000	2.676
7-8	4	1.31743	3.480	4.585	0.000	0.000	-0.163
8-9	5	1.35702	3.580	4.858	0.000	0.000	1.947
10-11	6	0.96664	3.580	3.461	0.000	0.000	1.299
	Total :	9.88996		40.605	0.000	0.000	16.628
Notes:	Center of grav Center of grav	vity of lenses vity of total	s are referre system is re	d to the fi ferred to f	ront surface first surface	e of each ce.	element.

Example 2:

WEIGHT CALCULATION:

This example shows how to calculate the weight for systems containing (front-surface) mirrors. In

order to obtain reasonable weight figures, a center thickness and a specific gravity of the mirror material must be assigned to mirror surfaces. This is accomplished by the commands THM and SPG We restore (load) the Cassegrain telescope from the examples library \optix\examples\mirror\cassegrain.otx and assign the following thicknesses to primary and secondary mirror:

thm s1 10.0 thm s2 5.0

Note that mirror thicknesses are always given as positive values. Next, specific gravities  $\rho$  must be specified for the mirrors. For example,

spg s1 3.1 spg s2 2.5

which specifies  $\rho$  in  $g/cm^3$  units. Now that all relevant data are entered, the WEI command outputs weight and center of gravity.

WEIGHT	CALCULATION:						
Surf.	Element Number	Volume (cm^3)	Gravity (g/cm^3)	Weight (g)	Cente X	r of Grav Y	rity Z
1-2	1 (	349.23284 379.59602 c: -30.36318 c:	3.100 ircular, tra ircular, obs	1082.622 nsmit) truct)	0.000	0.000	3.812
2-3	2	13.46352	2.500	33.659	0.000	0.000	-2.731
	Total :	362.69636		1116.281	0.000	0.000	-12.279
Notes:	Center of grav Center of grav	ity of lenses ity of total	s are referr system is r	ed to the fr eferred to f	ont surface irst surfac	of each e.	element.

Since a central obstruction has been assigned to the primary mirror (surface 1), weight calculation also reports the weight of the solid (unobstructed) mirror and the fictitious weight corresponding to the central obstruction, which is subtracted from the weight of the solid mirror.

## 12.7 Maximum Incidence Angles

This option traces ray bundles through the optical system for a given range of fields and zoom positions. The output reports the maximum ray incidence/refraction angles and the mean (average) incidence/refraction angles for each surface. Because the analysis is based on a full aperture ray trace, accuracy of the results may be increased by increasing NRD (number of rays across diameter).

Knowing the range of ray incidence angles is often helpful for designing multilayer coatings appropriately matched to the optical use of surfaces.

MAXAOI [fk fij	Calculates the maximum angle of incidence on all opti-
zk zij]	cal surfaces for a given range of field numbers fij
	and zoom positions zij. A description of the output
	is given below. Related commands: AOI, AOR, NRD.

#### **Description of output:**

BAY INCIDENCE ANGLES:

Analys in the	is is based on a entrance pupil	a full-aperture for each field	ray trace with and zoom positio	32 x 32 rays n.
Averag intens	e values are gi ity in the entr	ven with conside ance pupil.	ration of unifor	m and apodized
All in	cidence angles	are given in deg	rees.	
Zoom P	ositions : 1	- 1		
Fields	: 1	- 1		
	Average(deg)	Average(deg)	Maximum(deg)	Surface comment
Sur	(uniform)	(apodized)		
1	0.00000	0.00000	0.00000	
2	2.87489	1.64474	4.37264	Lens 1
3	9.62708	5.50348	14.70824	
4	1.77709	1.01125	2.78751	Lens 2
5	8.90122	5.09164	13.55067	
6	6.74561	3.85643	10.30278	

The average incidence angles are calculated in two variants. The column labeled 'uniform' assumes that all rays within the pupil have identical intensity (i.e. uniform intensity distribution), whereas the values in the column labeled 'apodized' take pupil apodization into account. The latter is often specified in systems using laser beams with a Gaussian intensity profile across the aperture.

#### 12.8 Optimal Coating Indices for Gradient Index Surfaces

This option determines the optimal index of refraction to use when AR coating a gradient index lens (front and back surfaces). Particularly for steeper curvatures the refractive index may vary considerably (as this is the intention in the design process), however, some unique index must be determined for the coating substrate. A commonly accepted estimate is the index at 70% of the clear aperture. Another, probably better, approach is the area-weighted index value, which is calculated by

$$n = \frac{\sum_{i=1}^{k} n_i (r_i^2 - r_{i-1}^2)}{r_{max}^2}$$
(12.1)

Both cases are calculated and the indices at the surface vertex and the clear aperture are given in addition. The command syntax is

CIND sk [ape1 ape2]	Output refractive indices to be used for coating a gradient index surface sk within clear apertures ape1 and ape2 of front and rear surface respectively. If ape1 and ape2 are omitted, the currently set apertures are used. Example:
	cind s2 10 9 ! Calculate optimal refractive indices at 10mm clear aperture (front surface) and 9mm clear aperture
	(rear surface).

#### A typical output in the text window would be

Refractive index values for AR-coating of gradient index lenses: Wavelength : 0.58760

	Area	70%		full	Clear
Surf	weighted	aperture	on-axis	aperture	aperture
1	1.7062033	1.7071323	1.7173626	1.6962368	12.500
2	1.6816796	1.6816665	1.6815213	1.6818191	11.255

## **12.9** Surface Sag

Surface sag computes the sag at any point on any surface in the optical system. The command syntax is:

	Surface sag (z-component) at surface sk and surface coordinates
SAG sk x_height	x_height, y_height, measured from the surface vertex with-
y_height [?]	out regard to tilt and decentration.

## **12.10** User Defined Graphics (UGR)

In addition to graphics predefined by the program, graphics defined by the user can be created. These are two-dimensional plots of any variable parameter against any performance measure known to OpTaliX. Parameters and functions may be composed from any command, arithmetic expression, function or macro as it would be entered in the command line. For example, changing the lateral displacement of a fiber in a fiber coupling optics is accomplished by the command

FRY .001

which offsets the receiving fiber 1  $\mu m$  from the nominal chief ray intercept in the image plane. In an user defined graphics (UGR), this misalignment may become a variable parameter by simply writing 'fry'. The function depending on this parameter, can also be any part of a command sequence, for instance 'SPD f3', which is the rms spot diameter at field number 3.

Let us assume, we want a plot of the coupling efficiency vs. the fiber misalignment. The commands required to achieve this are:

```
UGR X 'fry' LIM -0.005 0.005 0.001
UGR Y 'cef' LIM 0 1.0
```

The first line defines the variable parameter 'fry' to be plotted at the X-axis, the second line defines the dependent function 'cef', which is plotted at the Y-axis. The values following the token LIM define the lower and upper plot limits for X- and Y-axis and the variable step respectively. That is essentially all what is needed to define a user defined graphics (UGR). We may also want to add axis labels and a title to the plot:

```
UGR TIT 'Coupling efficiency vs. fiber misalignment'
UGR XLAB 'fiber decenter'
UGR YLAB 'CEF'
```

The plot is created with the command

UGR go

Here is a summary of all commands related to UGR:

	Define a variable used in	n UGR. var_string is a string (enclosed		
	in apostrophes) containing the variable definition. LIM is optional.			
	If given the plot limits are explicitly specified. Omitting LIM scales			
	the X-axis automatically. For example,			
UCD V was stains [ITM	ugr x 'thi s4'	! Thickness at surface 4 is variable in		
vlow which ystopl		UGR.		
xiow xiligii xscepj	ugr x '\$myvar'	! Creates a user-defined variable to be		
		varied in UGR.		
	ugr x 'yde s3	! UGR-variable definition with explicit		
	11m 0 30 .5'	limits.		
	Define a function used i	n UGR. var_string is a string (enclosed		
	in apostrophes) containi	ng the variable definition. LIM is optional.		
	If given the plot limits a	re explicitly specified. Omitting LIM scales		
UGR Y func_string [LIM	the Y-axis automatically.	For example,		
ylow yhigh]	ugr y 'efl'	! Calculate EFL and plot it as function		
	uan u lofi lim	Value.		
		- 200 mm)		
	Title string displayed in user-defined graphics. title_string			
	should be enclosed in apostrophes if the string contains blank			
	characters, otherwise ap	Difference in the online of example,		
UGR TIT title_string	ugr tit 'My	es title		
	uar tit stuff	as une.		
	ugi cit stull	title		
	V label displayed in y	and defined grouphing and label at using		
	should be enclosed in	apostrophes if the string contains blank		
	characters otherwise and	apositophes in the string contains blank		
LICD VIAD	ugr ylab / Y	Plots 'X variable' (without apostro-		
x label string	variable'	phes) as X-label.		
A	ugr xlab	! Plots 'x-value' (without apostrophes)		
	x-value	as X-label.		
	V-label displayed in us	ser-defined graphics vlabel string		
	should be enclosed in	apostrophes if the string contains blank		
	characters, otherwise apostrophes can be omitted. For example			
UGR YLAB	ugr vlab 'spd ! Plots 'Y variable' (without apostro-			
y_label_string	f1'	phes) as Y-label.		
	ugr xlab spd	Plots 'y-value' (without apostrophes)		
		as Y-label.		
UGR LOG floor	Select logarithmic display.			

A more user-friendly way is from the menu  $TOOLS \rightarrow User Defined Graphics$ , which invokes a dialog box to enter all required parameters. Our example discussed above as well as the resulting plot would look like (Fig. 12.3 and Fig. 12.4),

Litle: Ucupling efficiency vs. fibe	misalignment	
X - plot axis		
Variable parameter:	min max	Step
fry	-0.0050 0.0050	0.0010
X - label		
x-decenter		
Function:	min max	1
Function: CEF Y - label CEF	min max 0.0000 1.0000	
Function: CEF Y - label CEF Plot style	min max 0.0000 1.0000	
Function: CEF Y - label [CEF] Plot style C Linear connection	min max 0.0000 1.0000	ve settings
Function: CEF Y - label CEF Plot style C Linear connection Spline interpolation	min max 0.0000 1.0000 Restore settings Sa	ve settings
Function: CEF Y - label CEF Plot style C Linear connection Spline interpolation C Akima interpolation	min max 0.0000 1.0000 Restore settings Sa	ve settings

Figure 12.3: Dialog box to create an user defined graphics.

The string fields for the variable parameter and the function can be edited and expanded within the syntax rules given for each command. There are a limited number of predefined variables and functions, which may be accessed by clicking on the associated down arrows. A concise descriptive text is given to each variable/function string, separated by an exclamation mark "!". Text after the exclamation mark is considered as a comment and will thus be ignored. It is not part of the variable/function definition.

UGR definitions may be saved or restored (loaded) to/from a macro file with extension \*.ugr.

Due to the numerous number of plots which can be created with user defined graphics, there are no intelligent defaults for the independent variables or the dependent functions. In case of uncertainty, it is advisable to test the commands and the resulting function values in the command line prior to using them in the UGR option.

Also note, that some variables only work if the corresponding system parameter are properly defined. For example, a variable decenter (XDE or YDE) requires that the surface can be decentered (add "D" to surface type if needed).

#### 12.10.1 Variable Parameters in User-defined Graphics

Variable parameters in user-defined graphics (UGR) can be specified as follows:

• Any construction parameter that can be entered/edited on the command line can be made variable in UGR. For example, THI s4 (thickness at surface 4). Enter the parameter plainly, without quotes or apostrophes.

Variable parameter:	
THI s4	•

Specify any construction parameter as variable in UGR, just as you would enter it in the command line or in a macro.



Figure 12.4: Example output of user defined graphics: CEF vs. fiber misalignment.

• Specify any valid user-defined variable. Note for brevity: User-defined variables *must* begin with a "\$" character followed by at least one alpha-numerical character.

Variable parameter:	
\$var1	•

Enter a user-defined variable directly. The variable need not exist before, it is created during UGR execution.

#### 12.10.2 Functions and Macros in User-defined Graphics

In user-defined graphics (UGR), the function values to be plotted on the Y-axis of a graph can be defined by various methods:

• A lens database item (LDI) provides the easiest access to a lens construction parameter. See for example Fig. 12.3 which asks for coupling efficiency (CEF). Enter the name of this parameter enclosed in square brackets in the function field. For example,

Specify a lens database item (LDI) directly. In this example, the function value is the "equivalent focal length" (EFL).

• Specify an arithmetic expression which may include variables and lens database items (LDI).

Define an arithmetic expression, including a LDI.

• Specify a function which must have been previously defined in a separate command or a macro. For example, if we have defined the function "myfunc ==  $\$x^2$ " (without the quotes), the square of variable x would be returned.

Use a function previously defined for calculating the function value.

• Specify a macro which returns a value. In macros, (function-) values can be passed to the calling module using the RETURN statement (see page 474).

Run a macro which evaluates and returns the function value. See also RETURN (page 474), and RUN (page 458). The macro file is assumed in the macro directory as defined in the preferences settings (page 23) which is typically c:\programs\optalix\macro. For any different location you must explicitly specify the path.

#### 12.10.3 UGR Command Example

In addition to the menu-based entry of user-defined parameters, as described in the previous sections, this section gives a concise overview on defining user-defined graphics from the command line respectively from macros.

ugr X 'thi s2' LIM 0.5 1.0 0.05	Define the independent parameter (variable) range for UGR-plot. The variable parameter in this case is 'THI s2', thickness at surface 2. The variable parameter (thi s2) is varied within the limits 0.5 to 0.1 at steps of 0.05.
ugr Y 'spd f1 w1' LIM 0 0.1	Specify the dependent parameter (i.e. func- tion value). In this case the spot diameter at field 1, wavelength 1, (spd f1 w1) shall be cal- culated. The plot limits (i.e. along the Y-axis) are between 0.0 and 0.1. Note that these limits may change according to the parameter and functions defined.

ugr tit 'My UGR Graphics'

## 12.11 Analytical Setup

A few optical systems may be created from scratch by entering a few basic system parameters like focal length, aperture, field of view, etc. They are then automatically generated on the basis of thirdorder theory. This means, that the aberrations of the resulting systems are corrected to third order, neglecting any higher order aberrations. However, these systems provide a good starting point for further refinement or as building blocks to construct more complex systems.

#### 12.11.1 Lens of best Form

Constructs a lens of best form, for which the third-order spherical aberration reaches a minimum for a given object distance s and power  $\varphi$ . Without reiterating third-order theory, we first define auxiliary variables

$$A = \frac{2n+1}{n-1}, \qquad B = \frac{n+1}{n}, \qquad C = \frac{n+2}{n}$$
(12.2)

The curvatures of the lens are then obtained by

$$c_1 = \frac{A\varphi + 4B \cdot \frac{1}{s}}{2C}\varphi \tag{12.3}$$

$$c_2 = \left(c_1 - \frac{1}{n-1}\right)\varphi\tag{12.4}$$

#### **Command Syntax:**

SETUP SLE	Single lens setup. The lens bending is chosen to minimizing third-
	order spherical aberration. This command invokes a dialog box.

#### 12.11.2 Achromatic Doublet

Constructs a thin-lens achromatic doublet from selected materials and a given focal length. The algorithm is found in Laikin [29].

#### **Command Syntax:**

SETUP ACR	Thin-lens achromatic doublet setup. This command invokes a dialog
	box.

#### 12.11.3 Lurie-Houghton Telescope

Constructs a catadioptric telescope of Luri-Houghton form. The "Lurie-Houghton" telescope combines design elements from Lurie's original proposal [31] (two-lens full-aperture corrector) with elements of the Houghton telescope [21] (spherical corrector). Both modifications greatly simplify manufacturing, however, at the expense of astigmatism. A distinct advantage of this design form is the improved correction of coma compared to other catadioptric telescopes (Schmidt-Newton, Wright). A design example of the Lurie-Houghton design form can be found in the /examples/catadiop directory.

Analytical setup of the Lurie-Houghton design form is accomplished by a few simple equations. From the auxiliary variables

$$A = \frac{n+2}{n(n-1)^2}, \qquad B = \frac{2(2n+1)}{(n-1)^2}, \qquad C = \frac{2(n+1)}{n(n-1)}$$
(12.5)

$$D = d \cdot \varphi, \qquad L = \frac{(D-2)(2A-B)}{C}, \qquad Q = \frac{(2-D)L^2}{2C}$$
 (12.6)

we obtain the radii of the corrector

$$r_1 = -r_3 = \frac{2L(n-1)}{(Q+1)\varphi} \tag{12.7}$$



Figure 12.5: Lurie-Houghton design form.

$$r_2 = -r_4 = \frac{2L(n-1)}{(Q-1)\varphi}$$
(12.8)

with

- $\varphi$  optical power of the primary mirror =  $2/r_m$
- d distance of last corrector surface to primary mirror

#### **Command Syntax:**

SETUP LURIE	Setup of a Lurie-Houghton Telescope. A dialog box is invoked
	Setup of a Larie Houghton Telescope. A datiog box is invoked.

#### 12.11.4 Reflecting Telescopes

This section describes the theory for the setup of basic reflective telescopes (e.g. Parabola, Cassegrain, Gregory, Ritchey-Chretien, etc.).



Figure 12.6: Paraxial quantities at a compound telescope

#### **Command Syntax:**

SETUP TEL	Setup of compound reflecting telescopes such as Cassegrain, Richey- Chretien, Gregory or Parabola. A dialog box is invoked, which allows selection of the various design forms.
-----------	---------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------

The equations and formulae presented hereafter are deduced from R.N.Wilson [61]. The variables as shown in Fig. 12.6 are defined as

- $d_1$  Separation of primary mirror and secondary mirror
- *L* Distance of focus from secondary mirror
- *BF* Back focus (distance of focus from primary mirror)
- $f_1$  Primary mirror focal length
- $f_2$  Secondary mirror focal length
- $m_2$  Secondary mirror magnification

Note, that the sign convention is in accordance with the definitions given in chapter 2.

#### 12.11.4.1 Classical Cassegrain and Gregory Form

These forms are defined by a primary mirror of parabolic form  $(K_1 = -1)$ . The position of the secondary mirror is defined by:

$$d_1 = \frac{m_2 f_1 + BF}{1 - m_2} \tag{12.9}$$

The power  $\Phi_2$  of the secondary mirror is:

$$\Phi_2 = \frac{1}{f_2} = \frac{1}{BF - d_1} - \frac{1}{f_1 - d_1}$$
(12.10)

The conic constant of the secondary mirror is then a function of the secondary mirror magnification  $m_2$ :

$$K_2 = -\left(\frac{m_2 - 1}{m_2 + 1}\right)^2 \tag{12.11}$$

#### 12.11.4.2 The Aplanatic Telescope and its Ritchey-Chretien Form

The Ritchey-Chretien (RC) form is an important modification of the Cassegrain telescope. The RCsolution solves for the field coma of a 2-mirror telescope, which is zero for an aplanatic condition. The solution of the aspheric conic constants is achieved by:

$$K_1 = -1 + \frac{2L}{d_1 m_2^3} \tag{12.12}$$

$$K_2 = -\left[\left(\frac{m_2 - 1}{m_2 + 1}\right)^2 + \frac{2f'}{d_1 \left(m_2 + 1\right)^3}\right]$$
(12.13)

The power of the secondary mirror  $M_2$  is obtained from Eq. 12.10.

## 12.12 Slider Control

Sliders are used to interactively change any system or surface parameter. The result on system layout or performance can be immediately viewed in any analysis window. That is, the effect of changing values in the prescription of an optical system is immediately displayed in open analysis windows.

Sliders are invoked by the command SLID or from the main menu *Tools - Sliders*. A a dialog showing up to five slider controls is displayed (see Fig. 12.7).

📢 Slic	ler					_ 🗆 🗙
On	Construction Parameter	SUR/FLD/WL	Range min.	Range max.		Value
	CUY	S1 💌	-0.02000	0.04000		0.00880
	YAN	F2 💌	0.00000	10.00000		1.00000
◄	K	S1 💌	-1.00000	1.00000		-0.76000
	<b>_</b>	•	0.00000	0.00000		0.00000
	•	•	0.00000	0.00000		0.00000
	Save with prescription d	ata	Restore	Help	Close	

Figure 12.7: Slider Dialog. Allows definition of arbitrary construction parameters to be adjusted interactively while immediately viewing the analysis result in open windows.

Description of slider controls:

On	Turns on/off a specific control.
Construction Parameter	This is any construction or system parameter which can be entered in the command line. The pull-down menu offers a selection of pre- defined (mostly used) parameters, however, individual parameters can be entered in the first menu item (initially blank).
SUR/FLD/WL	This field expects a surface, field or wavelength qualifier such as $S3$ , $F2$ , or $W4$ . The allowable range of surface/field/wavelength qualifiers in the current optical system may be selected from the pull down menu.
Range min.	The minimum allowable value of a construction or system parameter.
Range max.	The maximum allowable value of a construction or system parameter.

#### Notes:

- Changes made to slider controls are immediately reflected in the surface editor. However, changes made in the surface editor directly (for example inserting or deleting surfaces) will not be updated in the slider dialog. If the optical system is changed, you are requested to close and reopen the slider dialog to update for the new parameters.
- Analysis windows that require long computing times (such as MTF, PSF, etc) may slow down window update significantly. If necessary, close computing intensive analysis windows.
- A copy is made of the data to be modified prior to displaying the slider dialog. The "Restore" button then restores the state of the optical system before the slider dialog was invoked.
- Slider settings can be saved with the current system by checking the "*save with prescription data*" check box found in the lower left corner of the dialog. This also implies that slider settings are specific to the current system.
- On closing the slider control dialog, the current slider settings are used for all subsequent analyses. Click on the "Restore" button before leaving the slider dialog if you want to return to the previous system (i.e. before the slider dialog has been invoked).

## 12.13 ECHO Command Line

ECHO Y N	Echoes commands (entered in the command line) in the text output window.
	Enabled by "Y" and disabled by "N". The default setting is "ECHO N". The
	ECHO command is only active for a particular session of $OpTaliX$ . ECHO
	does not apply to commands executed within a macro. If you want to disable
	all text output, use the "OUT SILENT" option (page 454).

## 12.14 CLS (Clear Screen)

	Clears the contents of the text window ("clear screen"). For Code V com- patibility, the CLS command can also be used for defining plot colours. See
CLS	sections
	7.2 (page 47) for defining field colours,
	20.1 (page 390) for defining coating colours.

## 12.15 Time

TIM	Outputs an	character	string	with	the	current	time	in	24	hour	format
	HH:MM:SS										

## 12.16 Date

DAT	Outputs an character string with the current date in the format DD MMMM YYYY.
-----	-------------------------------------------------------------------------------

## 12.17 File Name

FNAME	Outputs a character string containing the file name (without path).
FPNAME	Outputs a character string containing the file path + name

## 12.18 File Path

FPATH	Outputs an character string containing the file path only.	
# 12.19 Operating System Command

	Opens a command window (DOS-box) to exe-
	cute operating system (OS) commands. Con-
	trol is then transferred to the operating system
	and $OpTaliX$ waits until the OS command win-
	dow is closed (terminated). Under Windows
	95/98/Me operating systems command.com is in-
	voked. Windows NT/2000/XP operating systems
SYS [ 'cmd_string'   ? ]	call cmd.exe by default. The optional param-
	eter cmd_string is the operating system com-
	mand. It must be enclosed in apostrophes. The
	question mark "?" keeps the OS command window
	open, while omission of the question mark executes
	cmd_string in silent mode, except where SYS is
	given without any parameters.

#### **Examples:**

SYS	invokes (without control t	an OS comm the apostrop o OpTaliX.	hand window. The window remains open. Type 'exit' bhes) to close the OS command window and give back
SYS	'dir *.*' ?	invokes 'dir *.*' (without give bac	an OS command window, executes the system command and waits for additional OS commands. Type 'exit' t the apostrophes) to close the OS command window and k control to OpTaliX.
SYS	'copy a.txt	b.txt′	executes the OS command and gives back control to $OpTaliX$ immediately.

Note that operating system commands may also be used in macros where the form without the question mark "?" is preferable to ensure uninterrupted execution.

# 12.20 Logging Ray Data

It is sometimes desirable to have access to ray data, in particular if a large number of rays is concerned (such as in spot diagrams or in illumination calculations). Ray data can then be logged (written) to a file for later reuse.

RAYLOG sk off FIL log_file	surface sk to a file log_file. Specification of surface sk at which ray data are to be logged is mandatory. If omitted, the command is ignored. The "off" option or s0 disables ray logging. Ray data are written to plain ASCII files without header. See sect. 32.13 for a description of the ray file format. Examples: raylog s4 fil rays.txt ! logs all rays
	calculated in subsequent commands.
	raylog off ! disables ray logging.

Use this command with great care! There are many analysis options (such as PSF, MTF, spot and illumination calculations) which generate a massive amount of ray data and therefore log-files may become huge. Also do not forget to disable ray logging by the "RAYLOG off" command after you have acquired ray data. Otherwise rays may be inadvertently written to the file, thus using excess hard disc space and slowing down calculations due to hard disc writing.

The RAYLOG command is favorably used in a macro environment. For example, consider the following situation where ray data resulting from an illumination calculation at the image surface (the target surface) are stored in a file:

raylog si fil my_rays.txt	!	turn on ray logging
ill ?	!	invokes illumination dialog for editing
		illumination parameters
raylog off	!	turn off ray logging

With the example above, the ray data are then found in the file my\_rays.txt. See also sect. 32.13 (page 525) for a description of the ray file format.

# Materials, Glasses

13

A large number of optical materials is available in OpTaliX. The optical and physical constants of refractive materials are stored in several catalogue files. The currently available catalogues are:

Identifier	Manufacturer
SCH	Schott, 2000 catalogue
SCO	Schott, old catalogue
OHA	Ohara
COR	Corning
SUM	Sumita
HIK	Hikari
HOY	Ноуа
CAR	Cargille liquids
APE	Apel series from Mitsui Chemicals
CDG	CDGM Glass Co.
EPS	EP series
LPT	LightPath, axial gradients
NHG	HuBei New HuaGuang Information Materials
SEL	NSG, Selfoc <sup><math>TM</math></sup> radial gradients
GEL	Geltec
GLC	Gradient Lens Corp.
GRT	Grintech, Jena
ARC	Archer OpTx
OGC	Osaka Gas Chemicals
RPO	Rochester Precision Optics
RUS	Russian glass catalogue
SPE	Special materials (infrared, UV, plastic materials, liquids)
OBS	All obsolete materials from various vendors

The optical materials can be homogeneous or inhomogeneous in their refractive index. Standard materials from different suppliers are available in the spectral range from 200nm to  $30\mu$ m. Besides the refractive index information, a large number of additional optical and physical properties are provided:

- · Partial dispersion
- Linear expansion coefficient

- Transformation and melting temperature
- Thermal conductivity
- Specific weight
- Hardness
- E-Module
- Chemical properties
- Temperature coefficient of refractive index
- Internal transmission

Most of these data can be viewed and partly edited in the glass manager (see section 24, page 439). **Command Summary:** 

GLA [sij] [zij zk] [man:]glass_name	Glass name of manufacturer (e.g. BK7). man is optional and designates the manufacturer. The glass vendor may also be specified by preceding the glass name with the manufacturers short code followed by a colon, such as SCH:BK7. The length of the glass name, including the manufacturers short code is limited to 64 characters. See also section 13.3 for a list of manufacturers short codes.
GL1 [sij] gl1_name	Glass in front of surface (gl1_name is identical to GLA in classical (i.e. sequential) systems.
GL2 [sij] gl2_name	Glass at rear of surface (required for non-sequential surfaces only )
AIR [sij]	Medium is air
REFL [sij]	Medium is reflecting (mirror)
REFR [sij]	Medium is refracting (lens)
RMD [sij] REFR REFL TIR	Refractive/reflective mode. Available modes are REFR = refract all rays at surface(s) sij = default mode. REFL = reflect all rays at surface(s) sij TIR = only reflect rays that fulfil TIR condition This command complements the REFR, REFL and TIR com- mands.
IND [sij   wij] val_1 val_2 val_n	Refractive index (ordinary) corresponding to defined wavelengths. See also wavelength definition on page 48. Only takes effect for private glasses (see section 13.5). Examples: ind s3 1.541 1.540 1.490 ! defines indices for the first three wavelengths ind s3 w2 1.540 ! defines index at wavelength number 2.
	commuted on next page

continued from previous page		
INE [sij] val_1	Refractive index (extraordinary) for defined wavelengths	
val_2 val_n		
DVO [sij] delta_nue	Dispersion shift $\Delta \nu$ (in absolute $\nu$ -values). Example: DVO s35 4.2. See also section 13.1.12 for definition of the primary dispersion.	
DNO [sij] delta_n	Index shift $\Delta n$ at reference wavelength. Note: Reference wavelength is defined by REF command.	
PGO [sij]		
delta_P(g,F)	Offset of partial dispersion $P_{g,F}$ from catalogue value (see section 13.1.13 for definition of $P_{g,F}$ ).	
PCO [sij]		
delta_P(C,s)	Offset of partial dispersion $P_{C,s}$ from catalogue value (see sec-	
	tion 13.1.13 for definition of $P_{C,s}$ ).	

## 13.1 Dispersion

Dispersion describes the variation of the index of refraction as a function of wavelength. It is one of the most important factors in selecting optical materials. The "old Schott" formula and the Sellmeier formula are consistently used. The coefficients are stored in glass catalogue files, which requires only specification of the glass name. The correct indices of refraction are calculated from the coefficients for all specified wavelengths.

#### 13.1.1 Old Schott (Laurent) Formula

Formerly, Schott described the index of refraction in the visible portion of the spectrum by a Laurent series, sometimes called the "Schott formula"

$$n^{2}(\lambda) = A_{0} + A_{1} \cdot \lambda^{2} + A_{2} \cdot \lambda^{-2} + A_{3} \cdot \lambda^{-4} + A_{4} \cdot \lambda^{-6} + A_{5} \cdot \lambda^{-8}$$
(13.1)

where  $\lambda$  = wavelength in  $\mu$ m and n = refractive index.

#### 13.1.2 Sellmeier Formula

The Sellmeier formula has recently been adopted by Schott and other glass manufacturers.

$$n^{2}(\lambda) - 1 = \frac{B_{1}\lambda^{2}}{\lambda^{2} - C_{1}} + \frac{B_{2}\lambda^{2}}{\lambda^{2} - C_{2}} + \frac{B_{3}\lambda^{2}}{\lambda^{2} - C_{3}}$$
(13.2)

where  $\lambda$  = wavelength in  $\mu$ m.

#### 13.1.3 Extended Sellmeier Formulas

There are two forms to extend the standard Sellmeier formula as given in eq. 13.2 by adding more coefficients:

Sellmeier 3:

$$n^{2}(\lambda) - 1 = \frac{B_{1}\lambda^{2}}{\lambda^{2} - C_{1}} + \frac{B_{2}\lambda^{2}}{\lambda^{2} - C_{2}} + \frac{B_{3}\lambda^{2}}{\lambda^{2} - C_{3}} + \frac{B_{4}\lambda^{2}}{\lambda^{2} - C_{4}}$$
(13.3)

Sellmeier 5:

$$n^{2}(\lambda) - 1 = \frac{B_{1}\lambda^{2}}{\lambda^{2} - C_{1}} + \frac{B_{2}\lambda^{2}}{\lambda^{2} - C_{2}} + \frac{B_{3}\lambda^{2}}{\lambda^{2} - C_{3}} + \frac{B_{4}\lambda^{2}}{\lambda^{2} - C_{4}} + \frac{B_{5}\lambda^{2}}{\lambda^{2} - C_{5}}$$
(13.4)

where  $\lambda$  = wavelength in  $\mu$ m.

#### 13.1.4 Reduced Sellmeier Formulas

Sellmeier 2:

$$n^{2}(\lambda) - 1 = A + \frac{B_{1}\lambda^{2}}{\lambda^{2} - C_{1}} + \frac{B_{2}}{\lambda^{2} - C_{2}}$$
(13.5)

Sellmeier 4:

$$n^{2}(\lambda) = A + \frac{B_{1}\lambda^{2}}{\lambda^{2} - C_{1}} + \frac{B_{2}\lambda^{2}}{\lambda^{2} - C_{2}}$$
(13.6)

where  $\lambda$  = wavelength in  $\mu$ m.

#### 13.1.5 Nikon Dispersion Formula

This form is used by Nikon:

$$n^{2}(\lambda) = A_{0} + A_{1} \cdot \lambda^{2} + A_{2} \cdot \lambda^{4} + A_{3} \cdot \lambda^{-2} + A_{4} \cdot \lambda^{-4} + A_{5} \cdot \lambda^{-6} + A_{6} \cdot \lambda^{-8} + A_{7} \cdot \lambda^{-10} + A_{8} \cdot \lambda^{-12}$$
(13.7)

where  $\lambda$  = wavelength in  $\mu$ m.

#### 13.1.6 Herzberger Formula

The Herzberger equation combines Sellmeier and power series terms. It was first developed for glasses and later applied to infrared crystalline materials.

$$n = A + \frac{B}{(\lambda^2 - \lambda_0^2)} + \frac{C}{(\lambda^2 - \lambda_0^2)^2} + D\lambda^2 + E\lambda^4 + F\lambda^6$$
(13.8)

where the choice of the constant  $\lambda_0^2 = 0.028$  is arbitrary in that it is applied to all materials. The wavelength  $\lambda$  is given in  $\mu$ m.

#### 13.1.7 Hartmann Formula

$$n = A_0 + \frac{A_1}{(A_2 - \lambda)^{1.2}} \tag{13.9}$$

The wavelength  $\lambda$  is given in  $\mu$ m.

#### 13.1.8 Cauchy Formula

$$n = A_0 + \frac{A_1}{\lambda^2} + \frac{A_2}{\lambda^4} \tag{13.10}$$

The wavelength  $\lambda$  is given in  $\mu$ m.

#### 13.1.9 Conrady Formula

$$n = n_0 + \frac{A_1}{\lambda} + \frac{A_2}{\lambda^{3.5}} \tag{13.11}$$

The wavelength  $\lambda$  is given in  $\mu$ m.

#### 13.1.10 Handbook of Optics 1 Formula

$$n^{2} = A_{0} + \frac{A_{1}}{(\lambda^{2} - A_{2})} - A_{3}\lambda^{2}$$
(13.12)

The wavelength  $\lambda$  is given in  $\mu$ m.

#### 13.1.11 Handbook of Optics 2 Formula

$$n^{2} = A_{0} + \frac{A_{1} + \lambda^{2}}{(\lambda^{2} - A_{2})} - A_{3}\lambda^{2}$$
(13.13)

The wavelength  $\lambda$  is given in  $\mu$ m.

#### 13.1.12 Primary Dispersion

The difference in the refractive indices at the wavelengths corresponding to the F and C lines referred to the wavelength at the d-line is called the *primary dispersion*. It is expressed by the Abbe number

$$\nu = \frac{n_d - 1}{n_F - n_C} \tag{13.14}$$

where  $n_d$  is the index of refraction at 0.5876 $\mu m$ ,  $n_F$  is the index of refraction at 0.4861 $\mu m$  and  $n_C$  is the index of refraction at 0.6563 $\mu m$ .

#### 13.1.13 Partial Dispersion

The partial dispersion is expressed as the ratio

$$P_{x,y} = \frac{n_x - n_y}{n_F - n_C}$$
(13.15)

for two selected wavelengths x and y. In OpTaliX, the two commonly used partial dispersions in the visible and near-infrared portion of the spectrum are

$$P_{g,F} = \frac{n_g - n_F}{n_F - n_C} , \qquad P_{C,s} = \frac{n_C - n_s}{n_F - n_C}$$
(13.16)

# 13.2 dn/dT

The basic Schott model is used for the absolute index change from the index at standard temperature and pressure. It is given by

$$\frac{dn_{abs}(\lambda,T)}{dT} = \frac{n^2(\lambda,T_0)-1}{2\cdot n(\lambda,T_0)} \cdot \left(D_0 + 2\cdot D_1 \cdot \bigtriangleup T + 3\cdot D_2 \cdot \bigtriangleup T^2 + \frac{E_0 + 2\cdot E_1 \cdot \bigtriangleup T}{\lambda^2 - \lambda_{TK}^2}\right)$$
(13.17)

with:

 $T_0 = \text{Reference temperature (} 20^\circ\text{C}\text{)}$   $T = \text{Temperature (in }^\circ\text{C}\text{)}$   $\Delta T = \text{Temperature difference versus } T_0$  $\lambda = \text{Wavelength (in } \mu\text{m) in vacuum}$ 

 $\lambda_{TK}$  = average resonance wavelength (in  $\mu$ m)

Note that some glass manufacturers only provide dn/dT-data at discrete points (wavelengths and/or temperatures). In such cases, the data is fitted according to Eq. 13.2 in order to give a continuous representation of dn/dT. This may result in small (practically negligible) deviations from catalogue data in temperature calculations, when listing dn/dT (DNDT) data (see LIS DNDT command, page 179) or querying DNDT as lens database item (page 477).

# 13.3 Pre-defined Glass Catalogues

Glasses from glass manufacturers are designated on surfaces by an alphanumeric code. This code (a character string) may contain the glass name as well as the manufacturer short code (a 3 character string). If both, manufacturer short code and glass name are provided, they are separated by a colon. The general syntax is:

gla si..j [manuf:]name

An alphanumeric code, limited to 64 characters, from a manufacturers catalogue is entered.

#### **Examples:**

```
gla s1..3 BK7
gla s4 lak9
gla s2 sch:bk7
```

The manufacturers short codes are derived from the first 3 characters of the manufacturers name, which are given in table 13.2.

Table 13.2. Short codes of glass manufacturers		
Short Code	Glass Manufacturer	
SCH	Schott 2000	
SCO	Schott (old catalogue)	
OHA	Ohara	
HOY	Ноуа	
COR	Corning	
SUM	Sumita	
CAR	Cargille (liquids)	
LPT	LightPath (Gradium glass)	
GRT	GrinTech, Jena, gradient index glass	
NSG	Nippon Sheet Glass Company	
GLC	Gradient Lens Corp.	
CHI	Chinese catalogue	
	continued on next page	

Fable 13.2: Short cod	es of glass	manufacturers
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continued from previous page		
ARC	Archer OpTx	
SPE	Special Materials (Infrared, plastics, etc.)	

Glass name and manufacturer short code are case insensitive, e.g. BK7 and bk7 are treated as identical glasses.

# **13.4** User-defined (external) Glass Catalogues

OpTaliX provides the ability to convert external glass catalogues to a format which is used by OpTaliX. Currently the Zemax glass catalogues (extension .agf) can be converted to the OpTaliX format (extension .csv). The command to convert a glass catalogue is given in table 13.4:

CONVAGF agf_filename csv_filename vendor_string		
	Converts a glass catalogue in Zemax AGF format to an OpTaliX CSV	
	format. If necessary, the full path information must be provided. In-	
	clude the file specification in apostrophes if it contains blank charac-	
	ters. The parameter vendor_string is a character string of min-	
imum 3 characters and identifies the vendor (like SCH for Schot		
	OHA for Ohara, etc.).	
CONVAGE ?	As above, converts an AGF glass catalogue. The question mark "?"	
	invokes a dialog box for interactive editing of the file names.	

Table 13.3: Commands for converting AGF glass catalogues.

The converted glass catalogue (in OpTaliX CSV format) must be stored in the directory of USER Glass Catalogues. This is by default C:\ProgramData\OpTaliX\glasscat\. This directory can only be redefined in the preferences, see section 3.

**Warning:** Conversion of external glass catalogues can create conflicts with the built-in glass catalogues in OpTaliX and double entries of glass names may occur. To avoid this, the corresponding glass catalogue in OpTaliX can be deactivated. This can be accomplished in the main menue item Glass Manager --> Select Glass Catalogues, or by the command LOAD GCAT ?.

#### Example:

Converts the Zemax glass catalogue apel.agf to an OpTaliX glass catalogue apel.csv. The glass catalogue is denoted by the optional vendor string APEL.

convagf c:\temp\apel.agf c:\ProgramData\OpTaliX\glasscat\apel.csv APEL

# **13.5** Private Glasses

In most cases, the refractive index is implicitly defined by specification of a glass name. The refractive index is then calculated from coefficients stored in the glass catalogues. Other than the glass name, there is no further user interaction required to obtain the correct index. In some cases, however, it is necessary to explicitly enter the refractive index for given wavelengths, for example when exact coefficients are not available or to enter data for materials that are not included with OpTaliX.

With private glasses you enter your own glass names and associated index data. Private glasses are part of the lens in memory and only apply to that lens. Private glass data will be stored with the prescription data.

Private glasses must not be confused with melt glasses as described in the glass manager section 24.9, page 447. Melt glasses are also defined by wavelength/index pairs, however, they are stored in a separate glass catalogue file and are globally available within the OpTaliX environment.

Private glasses only retain to the current lens. To make private glasses available for use with several lenses, create a sequence (.SEQ file) with the desired private glass commands for all the glasses to be included and execute this sequence with each lens. A private glass must be defined before it can be specified on a surface.

Definition of private glasses can be accomplished in three ways,

- by entering pairs of wavelength and index of refraction, or
- by Laurent dispersion coefficients, or
- by glass manufacturers Sellmeier dispersion coefficients.

#### 13.5.1 Private Glass defined by Wavelength-Data Pairs

All private glass data are enclosed by the PRV, END commands. The example below shows definition of a private glass (mybk7) using wavelength-index data pairs:

PRV PWL 0.435 0.479 0.547 0.587 0.656 'myBK7' 1.527 1.523 1.519 1.5168 1.514 END

## 13.5.2 Private Glass defined by Laurent Dispersion Coefficients

Private glasses using Laurent coefficients are defined by entering the glass name, dispersion formula type and dispersion coefficients. The Laurent dispersion formula uses the LAU designator right to the glass name:

```
PRV
'myBK7' LAU AO A1 A2 A3 A4 A5
END
```

The sequence of the LAU coefficients is according to equation 13.1.

## 13.5.3 Private Glass defined by Sellmeier Dispersion Coefficients

The Sellmeier dispersion formula uses the GMS (glass manufacturers Sellmeier) designator right to the glass name:

```
PRV
'myBK7' GMS B1 C1 B2 C2 B3 C3
END
```

The sequence of the GMS coefficients is according to equation 13.2.

## 13.5.4 Private Glass defined by Hartmann Dispersion Coefficients

The Hartmann dispersion formula uses the HAR designator right to the glass name:

```
PRV
'myBK7' HAR A0 A1 A2
END
```

The sequence of the HAR coefficients is according to equation 13.9.

## 13.5.5 Private Glass defined by Cauchy Dispersion Coefficients

The Cauchy dispersion formula uses the CAU designator right to the glass name:

```
PRV
'myBK7' CAU AO A1 A2
END
```

The sequence of the CAU coefficients is according to equation 13.10.

These command sequences may also be conveniently stored in a macro file and then executed by the RUN command. The wavelength/index pairs need not to be sorted for (ascending or descending) wavelength. Wavelength values should be specified in micrometers (the default in OpTaliX), however, wavelengths in nanometer are also recognized to support compatibility with Code V syntax. Wavelength data > 100 are interpreted as nanometers (nm), otherwise micrometer ( $\mu m$ ) are assumed.

Private glasses may be specified on surfaces like any other catalogue glass, except that the glass name must be enclosed in apostrophes. Example:

gla s2 'MYBK7'

Also note that names given to private glasses are case sensitive, i.e. 'MYBK7' and 'mybk7' are treated as two separate glasses.

PRV	
	Start private glass entries. It accepts then PWL commands
	and 'glass_name' entries until terminated with and END
	command. Any other $OnTaliX$ command can be used
	within the DRV END environment See also the END
	command halow
	command below.
	Enter wavelength (in $\mu m$ ) for next refractive indices.
	This command is only required for wavelength-
	index data pairs. Up to 20 wavelengths are accepted.
	Wavelength data may also be entered in nanometers
	(nm) for Code V compatibility. Values $> 100$ are
	interpreted as nanometers, otherwise in micrometers
PWL wavel_1wavel_20	(μm).
	Private wavelength data should at least span the
	wavelengths to be used in calculations, as defined in
	the system data, or by the WL command. Interpola-
	tion will be done as necessary; extrapolation outside
	this range will be done, but accuracy is not assured.
	continued on next page
	]

continued from previous page					
'glass_name' index_1 index_20	For wavelength-index data pairs, enter up to 20 indices for the user-defined 'glass_name' with index values corresponding in order and number to the prior PWL com- mand. If 'glass_name' matches a catalogue glass, the catalogue glass always takes precedence, i.e. the private glass data will be ignored.				
'glass_name' LAU GMS HAR CAU coeff_1 coeff_6	For dispersion coefficients, enter up to 6 coefficients for the user-defined 'glass_name'. If 'glass_name' matches a catalogue glass, the catalogue glass always takes precedence, i.e. the private glass data will be ignored.				
END	Terminates entry of private glass data, started by PRV.				
IND sk [wk]	Returns index of refraction at surface sk and wavelength number wk in macros and lens database queries. Omission of wk returns the index at the reference wavelength. Note that IND may also be used for direct index specification (see obsolete commands below).				
Obsolete commands:					
IND sk sij index_1 index_11	Directly specify indices for the wavelengths currently in use (see WL command) without an underlying disper- sion model. That is, the indices entered on surface(s) sk sij must correspond to the system wavelengths. The obligatory glass name must be 'PRI' (without the apostrophes), see also next row. Although still available, use of this command is discouraged. Use the PRV - END construct as described in the commands above. The prob- lem with direct index specification arises if wavelengths are changed (for example using the WL command [page 48] or the EDI CNF command [page 44] via the configuration di- alog). In such cases the refractive index data assigned to the surfaces cannot be updated for glasses with direct index specification. It is therefore the users responsibility, to take care of this index to wavelength relation.				
GLA sk sij PRI	Defines a private glass with direct refractive index specifi- cation. The refractive indices must correspond to the sys- tem wavelengths and must be entered using the IND com- mand.				

## **General Notes on Private Glasses:**

Private glasses defined with the same name as an already existing private glass will change the data for the designated glass. Private glasses for which the glass name matches a catalogue glass, the catalogue glass always takes precedence, i.e the private glass data will be ignored.

Refracting indices for each system wavelength are fitted according to the old Schott formula (see Eq. 13.1).

# **13.6 Fictitious Glasses**

In contrast to the finite number of real glasses, fictitious glasses are defined in a continuous glass model, and in theory allow an infinite number of available glasses. The dispersion of fictitious glasses is defined internally, and is derived from the Abbe-number  $\nu$  and the partial dispersions  $P_{g,f}$  and  $P_{C,s}$ . Fictitious glasses are defined by two parameter:

- the refractive index  $n_d$  at the wavelength  $\lambda = 587.56nm$ ,
- the Abbe-number, which is a measure of the refractive index change with wavelength (  $\lambda = 486.13nm$  and  $\lambda = 656.27nm$ ) (see also section 13.1.12).

Fictitious glasses are denoted by a string of numeric digits of the following forms:

```
xxx.yyy where xxx = n_d - 1 and yyy = 10\nu_d
or: xxxyyy where xxx = n_d - 1 and yyy = 10\nu_d
```

The six-digit representation is also known as MIL-number. The length of the string is limited to 10 characters. Fictitious glasses are identified by the decimal point (anywhere within the string) or by the first character, which is a numeric digit. Consequently, a decimal point or a numeric digit as the first character is not allowed in any other glass codes. Since fictitious glasses are generic, properties other than refractive index and dispersion are not available. The fictitious glass model is restricted to the "visible" wavelength region, i.e. between 400nm and 700nm. Extension to shorter and larger wavelengths is only possible with reduced accuracy.

#### **Examples:**

GLA	s3	514.642	Define fictitious glass at surface 3 with $n_d$ 1.514 and $\nu_d = 64.2$				$d_d =$	
GLA	s3	514642	Define SCHOT	fictitious T code nur	glass nber (N	by 1IL-r	entering 1umber)	the

#### Notes:

- Fictitious (or MIL-number) glasses are an approximation to real glasses. According to its definition, fictitious glasses should only be used in the visible range. Outside the visible wavelength range (ultraviolet or infrared) the fictitious glass model is not accurate and should be avoided.
- Fictitious glasses may be automatically converted to the nearest (regular) catalogue glasses as described in section 12.4 on page 200.

# **13.7** Special Materials

"Special" materials are all materials like plastic, crystals, liquids, semi-conductors etc. Also the Schott Glass filters are found in the special catalogue. The data used in the SPECIAL catalogue are from various literature sources and data sheets of material manufacturers. Many of the data provided are relatively inaccurate or were not measured at sufficiently small spectral intervals, respectively there are systematic differences among the literature sources. Apart from the measurement uncertainties, many of the data were taken at temperatures other than 20°C. This may cause incorrect results if a system is analyzed at 20°C while the refractive index base is at another temperature. The user should be aware of it.

Material name	Spectral range $(\mu m)$	Description	Reference
AIR	0.2 - 15	Air	Kohlrauch [28], see also section 13.8 on page 236.
AGCL	0.5 -14	Silver Chloride	JOSA Vol.40, No.8, p.540
AGCL_IR	6.0 - 20.0	Silver Chloride, infrared band	JOSA Vol.40, No.8, p.540
ALON	0.4 - 2.3	Aluminum Oxynitride (ALON) Spinel	Handbook of Optics, Second Edi- tion, Vol2, 1995
AMTIR1	7.0 - 12.0	Ge <sub>33</sub> As <sub>12</sub> Se <sub>55</sub>	P.Klocek, Handbook of Infrared Optical Materials
AMTIR1A	1.5 - 12.0	$Ge_{33}As_{12}Se_{55}$	AmorphousMaterials,(www.amorphousmaterials.com)
AQUEOUS	0.36 - 1.1	Ocular medium	Navarro et.al., JOSA A, Vol2., No.8, pp.1274
AS2S3	1.0 - 9.0	Arsenic Sulfide	Handbook of Optics, 1978
B270	0.36 - 1.06	Desag float glass, super- white	Desag data sheet
BAF2	0.4 - 10.0	Barium Fluoride	JOSA Vol.40, No.8, p.540
BATIO3	0.4 - 0.7	Barium Titanate (BaTiO <sub>3</sub> )	Handbook of Optics, Second Edi- tion, Vol2, 1995
BGG	0.4 - 5.5	Barium Gallogermanate Glass	Appl. Opt., Vol.41, No.7, March 2002, pp. 1366
CAF2	0.42 - 5.0	Calcium Fluoride	Appl.Optics, Vol.2, No.11, p.1103
CAF2_IR	3.0 - 9.0	Calcium Fluoride, in- frared band	Appl.Optics, Vol.2, No.11, p.1103
CAF2_UV	0.15 - 2.0	Calcium Fluoride, ultravi- olet band	Schott Lithotec datasheet
CAF2_VIS	0.365 - 1.06	Calcium Fluoride, visible band, enhanced interpola- tion accuracy	Appl.Optics, Vol.2, No.11, p.1103
CERAM-Z	0.4 - 1.6	Clearceram-Z	Zero-expansion glass-ceramics, Ohara data sheet
CERAM- ZHS	0.4 - 1.6	Clearceram-Z HS	Zero-expansion glass-ceramics, Ohara data sheet
CDTE	1.0 - 30.3	Cadmium Telluride	Palik, Handbook of Optical Con- stants of Solids, Academic Press 1985
CLEARTRAN	0.45 - 10.0	"Cleartran" (water clear ZnS)	Rohm & Haas Advanced Materials data sheet (www.cvdmaterials.com)
COR9754	0.42 - 5.2	Germanate glass	Corning, France, data sheet
CORNEA	0.36 - 1.1	Ocular medium	Navarro et.al., JOSA A, Vol2., No.8, pp.1274
			continued on next page

# 13.7.1 Infra-red Materials, Plastics

continued from	previous page		
CSBR	0.5 - 22.0	Cesium Bromide	Journal of Research of the National
			Bureau of Standards, Vol. 51, No.3,
			1953, p.123
CSJ	0.3 - 26.0	Cesium Iodide	JOSA, Vol.45, No.11, p.987
CSJ_IR	9.0 - 40	Cesium Iodide	JOSA, Vol.45, No.11, p.987
DIAMOND	0.3 - 20	CVD-Diamond	Diamond Materials,
			www.diamond-materials.com
EYELENS	0.36 - 1.1	Ocular medium	Navarro et.al., JOSA A, Vol2.,
			No.8, pp.1274
GASIR1	2.0 - 14.0	Ge22As20Se58	Umicore technical data sheet
GASIR2	2.0 - 14.0	Ge22Sb15Se65	Umicore technical data sheet
GERMANIUN	1 2.99 - 13.2	Germanium, poly-	JOSA, Vol.48, Aug.1958, p.579,
		crystalline	Salzberg & Villa
GE_POLY	2.99 - 13.2	Germanium, poly-	JOSA, Vol.48, Aug.1958, p.579,
		crystalline	Salzberg & Villa
GE_MONO	2.9 - 22.0	Germanium, mono crys-	JOSA, Vol.48, Aug.1958, p.579,
		talline	Salzberg & Villa
HERASIL	0.22 - 2.3	Fused quartz	Heraeus datasheet
HOMOSIL	0.22 - 2.3	Fused quartz	Heraeus datasheet
INFRASIL	0.22 - 2.3	Fused quartz	Heraeus datasheet
IRG2	0.405 - 4.59	Chalcogenide glass	Schott datasheet
IRG3	0.656 - 4.59	Chalcogenide glass	Schott datasheet
IRG7	0.486 - 3.3	Chalcogenide glass	Schott datasheet
IRG9	0.404 - 3.3	Chalcogenide glass	Schott datasheet
IRGN6	0.486 - 3.3	Chalcogenide glass	Schott datasheet
IRG100	1.0 - 14.0	Chalcogenide glass	Schott datasheet
IRG11	0.58 - 4.59	Chalcogenide glass	Schott datasheet
IRTRAN1	1.1 - 6.2	MgF <sub>2</sub>	P.Klocek, Handbook of Infrared
			Optical Materials
KBR	0.5 - 12.0	Potassium Bromide	SPIE, Vol.400, p.141
KCL	0.5 - 12.0	Potassium Chloride	SPIE, Vol.400, p.141
KRS5	1.0-22.0	Thallium Bromoiodide	JOSA, Vol.46, No.11, p.956
LIF	0.19 - 5.5	Lithium Fluoride	The Infrared Handbook, IRIA,
			William L. Wolfe
LIF_IR	5.0 - 11.0	Lithium Fluoride, IR-	Handbuch der Physik
		band	
LIF_UV	0.19 - 1.2	Lithium Fluoride, UV-	Handbuch der Physik
		band	
LUMICERA	0.40 - 0.7	Lumicera, transparent ce-	Datasheet from Murata Manufac-
		ramics	turing Co. Ltd., 4-4-1 Higashi-
			Okino, Yokaichi city, Shiga 527-
			8558, Japan.
MACROLON	0.36 - 1.06	"Bayer" trade name	
MGF2	0.2 - 7.0	Magnesium Fluorite,	Appl.Optics, Vol.23, No.12, p.1980
		ordinary index, wide	
		spectral range, Sellmeter	
		equation	
			continued on next page

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MGF2_O	2.2 - 7.0	Magnesium Fluorite, or-	Appl.Optics, Vol.23, No.12, p.1980
MCE2 E	22.70	Magnasium Eluarita au	Appl Option Vol 22 No 12 p 1080
MGF2_E	2.2 - 7.0	magnesium Fluorite, ex-	Appl.Optics, vol.25, No.12, p.1980
MCE2 VO	0.2.2.0	traordinary index	A and Oction Met 22, No. 12, or 1000
MGF2_VO	0.2 - 3.0	Magnesium Fluoride	Appl.Optics, Vol.23, No.12, p.1980
MGO	0.5 - 5.1	Magnesium Oxide	E.D. Palik, Handbook of Optical
			Constants of Solids II
MGO_IR	2.5 - 5.55	Magnesium Oxide	E.D. Palik, Handbook of Optical
			Constants of Solids II
NACL	0.5 - 12.0	Natrium Chloride	
NOA61	0.36 - 2.3	Norland adhesive cement	Norland data sheet
PBF2	0.4 - 10.0	Lead Fluoride	
PMMA	0.36 -1.06	Polymethyl Methacrylate	Photonics design and applications
		(Lucite, Plexiglass)	handbook, 1996
POLYCARB	0.36 - 1.06	Polycarbonate (Lexan,	Germanow Simon Corp. datasheet
		Merlon)	*
OUARTZ	0.2 - 3.5	Fused quartz	equivalent to Suprasil, data from
		1	Heraeus datasheet
OUARTZ_IR	0.9 - 3.4	Fused quartz	Heraeus datasheet
SAPPHIRE	0.27 - 5.4	Sapphire	JOSA, Vol.52, No.12, p.1377
SILICA	02-35	Fused quartz (Suprasil)	Heraeus datasheet
SILICON	2 43 - 11 2	Silicon	Applied Optics Vol 19 No 24
SILICOI	2.45 11.2	Silicon	np $4130$ (1980) Salzberg & Villa
			data. It appears that these data are
			also used in Code V
	14.00	Silicon	Leade Ditcher data sheet
SILICON2	1.4 - 9.0	Silicon	Lulli Defrective Index of Sili
SILICONS	1.3 - 12.0	Shicon	H.H.LI, Refractive index of Sili-
			Length and Tenengentum Device
			length and Temperature Deriva-
			tives, J.Phys.Chem. Ref.Data,
	0.04 1.04		Vol.9, No.3, 1980
STYRENE	0.36 - 1.06	Polystyrene (Dylene, Sty-	Germanow Simon Corp. datasheet
		ron, Lustrex)	
SUPRASIL	0.27 - 3.5	tused quartz	Heraeus datasheet
TGG	0.38 - 1.6	Terbium Gallium Garnet	U.Schlarb, B. Sugg, "Refractive In-
			dex of Terbium Gallium Garnet",
			physica status solidi (b) 182, K91
			(1994)
TOPAS5013	0.4 - 1.07	Cyclic olefin copolymer	Ticona datasheet
		(COC)	
VACUUM	0.2 - 1.1	Vacuum	F.Kohlrauch, "Praktische Physik",
			1968, Vol.1, p.408
VITREOUS	0.36 - 1.1	Ocular medium	Navarro et.al., JOSA A, Vol2.,
			No.8, pp.1274
WATER	0.38 - 0.72	Water	
WATER2	0.40 - 0.80	Water with dn/dt data	R.C.Millard, G.Seaver [38]
SEAWATER	0.40 - 0.80	Seawater with dn/dt data	R.C.Millard, G.Seaver [38]
	1	1	continued on next page

continued from	previous page		
ZEONEX330	R 0.36 - 0.80	Cyclo Olefin Polymer	Zeon-Europe
ZEONEXE48	R 0.36 - 1.7	Cyclo Olefin Polymer	Zeon-Europe
ZEONEX480	R 0.40 - 1.0	Cyclo Olefin Polymer	Zeon-Europe
ZERODUR	0.4 - 0.7	Zerodur	Schott datasheet, and Schott TIE-43
			"Optical properties of Zerodur"
ZNS	0.4 - 0.8	Zink Sulphide, visible and	Morton datasheet
		medium infrared (Trade	
		name:Cleartran)	
ZNS_IR	3.0 - 12.0	Zink Sulphide, infrared	Morton datasheet
ZNS_M	0.4 - 8.0	Zink Sulphide, multispec-	Morton datasheet
		tral	
ZNS_M_IR	3.0 - 12.0	Zink Sulphide, multispec-	Morton datasheet
		tral	
ZNSE	0.54 - 10.2	Zink Selenide	Morton datasheet
ZNSE_IR	7.8 - 18.2	Zink Selenide, infrared	Morton datasheet

## **13.7.2** Schott Filter Glasses

BG3	FG03	GG385	KG01	NG01	OG515	RG09	UG01	VG06	WG225
BG4	FG13	GG395	KG02	NG03	OG530	RG610	UG05	VG09	WG280
BG7		GG400	KG03	NG04	OG550	RG630	UG11	VG14	WG295
BG12		GG420	KG04	NG05	OG570	RG645			WG305
BG18		GG435	KG05	NG09	OG590	RG665			WG320
BG20		GG455		NG10		RG695			
BG23		GG475		NG11		RG715			
BG24		GG495		NG12		RG780			
BG25						RG830			
BG26						RG850			
BG28						RG1000			
BG34									
BG36									
BG38									
BG39									
BG40									
BG42									

## 13.7.3 Schott Radiation Resistant Glasses

The impact of high energy photon- and particle radiation reduces the spectral transmission of optical glasses. For example, this effect can already be observed at Gamma radiation of  $10^3$  rad (1.25 MeV) as a browning of the glass. The intensity of this change in colour is not only a function of the type of radiation and its dose, it also depends on the energy of the ionizing radiation.

Doping glasses with  $CeO_2$  stabilizes them against colouring. Typically, the threshold at which colouring begins is raised to about  $10^6$  rad, at the expense of a reduced transmission in the blue.

The glass name of  $CeO_2$  doped glasses is appended with the letter "G" and a 2-digit number, indicating the amount of cerium oxide. For example, BaK1 G12 corresponds to 1.2% cerium oxide. Available radiation resistant glasses from Schott:

BK7G18	SSK5G06	BK7G25
LAK9G15	K5G20	LF5G15
BAK1G12	F2G12	SK4G13
SF5G10	SK5G06	SF6G05
SK10G10	SF8G07	KZFS4G20
GG375G34		

## 13.7.4 Gradient Index (GRIN) Glasses

The glass catalogues store gradient index materials with radial and axial index profile from Nippon Sheet Glass (NSG), Gradient Lens Corporation (GLC) and LightPath (LPT). The following materials are available:

Manufacturer	Code	Name	$z_{max}$	n(587nm)	Profile	Remarks/Product Code
LightPath	LPT	G14SFN	5.800	1.8049	axial	
LightPath	LPT	G14SFP	5.800	1.6489	axial	
LightPath	LPT	G22SFN	9.100	1.7860	axial	
LightPath	LPT	G22SFP	9.100	1.6569	axial	
LightPath	LPT	G23SFN	9.400	1.7758	axial	
LightPath	LPT	G23SFP	9.400	1.6561	axial	
LightPath	LPT	G32SFN	12.100	1.7666	axial	
LightPath	LPT	G32SFP	12.100	1.6731	axial	
LightPath	LPT	G41SFN	12.10	1.7443	axial	
LightPath	LPT	G41SFP	12.10	1.6961	axial	
LightPath	LPT	G51SFN	14.800	1.7446	axial	
LightPath	LPT	G51SFP	14.800	1.6982	axial	
LightPath	LPT	G4LAKN	13.931	1.7384	axial	
LightPath	LPT	G4LAKP	13.931	1.6726	axial	
NSG	SEL	SLN20	-	1.5845	radial	
NSG	SEL	SLS10	-	1.5477	radial	
NSG	SEL	SLS20	-	1.5477	radial	
NSG	SEL	SLW10	-	1.5868	radial	
NSG	SEL	SLW18	-	1.5868	radial	
NSG	SEL	SLW20	-	1.5868	radial	
NSG	SEL	SLW30	-	1.5868	radial	
NSG	SEL	SLH18	-	1.6294	radial	
NSG	SEL	SLA06	-	1.5238	radial	
NSG	SEL	SLA09	-	1.5845	radial	
NSG	SEL	SLA12	-	1.5930	radial	
NSG	SEL	SLA06A	-	1.5238	radial	
NSG	SEL	SLA09A	-	1.5845	radial	
NSG	SEL	SLA12A	-	1.5900	radial	
NSG	SEL	SLA20A	-	1.6098	radial	
Gradient Lens	GLC	EG10	-	1.5204	radial	
Gradient Lens	GLC	EG20	-	1.5204	radial	
Gradient Lens	GLC	EG27	-	1.5204	radial	
Gradient Lens	GLC	EG31	-	1.5204	radial	

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GrinTech rods	<b>GrinTech rods:</b> The GrinTech product code is represented in a short form. The number in the 'GT050',						
'GT100', or 'GT180' strings denotes the focal length (e.g. 050 = 0.5mm focal length), whereas the							
appendix denot	appendix denotes the intended wavelength: $06 = 670$ nm, $08 = 810$ nm, $13 = 1310$ nm, $15 = 1550$ nm.						
Grintech	GRT	GT050-06	-	1.62885	radial	GT-LFRL-050-025-50-CC (670nm)	
Grintech	GRT	GT100-06	-	1.62885	radial	GT-LFRL-100-025-50-CC (670nm)	
Grintech	GRT	GT180-06	-	1.62885	radial	GT-LFRL-180-025-50-CC (670nm)	
Grintech	GRT	GT050-08	-	1.623	radial	as above, at 810nm	
Grintech	GRT	GT100-08	-	1.623	radial	as above, at 810nm	
Grintech	GRT	GT180-08	-	1.623	radial	as above, at 810nm	
Grintech	GRT	GT050-13	-	1.616	radial	as above, at 1310nm	
Grintech	GRT	GT100-13	-	1.616	radial	as above, at 1310nm	
Grintech	GRT	GT180-13	-	1.616	radial	as above, at 1310nm	
Grintech	GRT	GT050-15	-	1.615	radial	as above, at 1550nm	
Grintech	GRT	GT100-15	-	1.615	radial	as above, at 1550nm	
Grintech	GRT	GT180-15	-	1.615	radial	as above, at 1550nm	
Grintech	GRT	GT100	-	1.530	radial		
Grintech	GRT	GT180	-	1.530	radial		
			-				
Grintech	GRC	GC050-06	-	1.524	cyl.	GT-LFCL-050-024-20 (670nm)	
Grintech	GRC	GC100-06	-	1.524	cyl.	GT-LFCL-100-024-20 (670nm)	
Grintech	GRC	GC130-06	-	1.524	cyl.	GT-LFCL-130-024-20 (670nm)	
Grintech	GRC	GC050-08	-	1.624	cyl.	GT-LFCL-050-024-50-CC (810)	
Grintech	GRC	GC100-08	-	1.624	cyl.	GT-LFCL-100-024-50-CC (810)	
Grintech	GRC	GC130-08	-	1.624	cyl.	GT-LFCL-130-024-50-CC (810)	
Grintech	GRC	GC050-09	-	1.621	cyl.	GT-LFCL-050-024-50-CC (940)	
Grintech	GRC	GC100-09	-	1.621	cyl.	GT-LFCL-050-024-50-CC (940)	
Grintech	GRC	GC130-09	-	1.621	cyl.	GT-LFCL-050-024-50-CC (940)	

#### 13.7.5 Liquids and Gels

A few specialty optical liquids from Cargille Laboratories Inc.[8] are stored in the glass database. They are grouped according to intended application as recommended by the manufacturer:

Immersion	:	Immersion liquids permit detection of imperfection in transparent and translucent materials and examination for stress and strain effects.						
Laser	:	High transmis	High transmission and highly stable liquids for laser wavelengths.					
EC-Series	:	High refractive	High refractive index, abnormal dispersion liquids. Low stability.					
E, H, M-Series	:	Ultra-high refractive index, toxic and corrosive.						
Matched	:	Matches precisely the refractive index of fused silica and closely approximates its dispersion.						
Gel	:	Optical coupla reflections or f	ant gel for op for mode stripp	otical fibers to reduce or eliminate internal ping.				
		Name	Application	$n_D(589.3nm)$ at 20.0°C				
			-					

Name	Application	$n_D(589.3nm)$ at 20.0°C
CG1050_1	Immersion	1.400
CG1050_2	Immersion	1.425
	·	continued on next page

continued on next page

continued from	m provious page							
	CC1050.3   Immersion   1.459							
CG1050_3	Immersion	1.458						
CG5040_4	Immersion	1.475						
CG5040_5	Immersion	1.500						
CG5040_6	Immersion	1.535						
CG5040_7	Immersion	1.570						
CG4550	Immersion	1.452						
CG433	Laser	1.295						
CG3421_1	Laser	1.320						
CG3421_2	Laser	1.400						
CG1056_1	Laser	1.400						
CG1056_2	Laser	1.455						
CG5610	Laser	1.475						
CG5763_1	Laser	1.600						
CG5763_2	Laser	1.630						
CGEC_164	<b>EC-Series</b>	1.640						
CGM_178	M-Series	1.780						
CGH_181	H-Series	1.810						
CGE_155	E-Series	1.550						
CG50350	Matched	1.4587						
CG06350	Matched	1.4587						
CG0607	Gel	1.457						
CG0608	Gel	1.457						

It is important to note that the index of refraction of liquids is highly dependent on temperature. Typically, the dn/dT values of liquids are about a factor of 100 larger than those of optical glasses. The dispersion coefficients stored in the glass catalogue are always based on 25.0°C.

# 13.8 Air, Vacuum

There are two predefined optical "materials", air and vacuum. Physically, the refractive index of air is  $n_{air} = 1.000273$  at normal temperature (20°C) and normal pressure ( $0.101325 \cdot 10^6$  Pascal). According to standard practice, however, the index of air is regarded to be 1.0, rather than its true value. This approach is justified because the vast majority of optical systems are designed and used under normal atmospheric conditions (sea level). In addition, all standard glass catalogues have indices expressed relative to 1.0. Only very few (specialized) designs are used in vacuum. Thus, when entering the medium "air", the refractive index is uniformly set to 1.000 for all specified wavelength. The index of air is altered by temperature and pressure in accordance with standard physical models. A good approximation, which also accounts for the wavelength dependence, is [28, 48]

$$n_{Air}(\lambda, T, p) = 1 + \frac{n_{Air}(\lambda, 15C, p_0) - 1}{1 + 3.4785 \cdot 10^{-3} \cdot (T - 15)} \cdot \frac{p}{p_0}$$
(13.18)

$$n_{Air}\left(\lambda, 15 degC, p_0\right) = 1 + \left\{ 6432.8 + \frac{2949810 \cdot \lambda^2}{146 \cdot \lambda^2 - 1} + \frac{25540 \cdot \lambda^2}{41 \cdot \lambda^2 - 1} \right\} \cdot 10^{-8}$$
(13.19)

with

- $p_0 = 0.101325 \cdot 10^6$  Pa (= normal pressure in Pascal)
- p = Pressure of air in Pascal
- $\lambda$  = Wavelength in  $\mu m$  in vacuum
- T = Temperature in °C

The temperature dependance of the index of air is given by [48]

$$\frac{dn_{Air}(\lambda,T)}{dT} = -0.00367 \cdot \frac{n_{Air}(\lambda,T,p) - 1}{1 + 0.00367 \cdot T}$$
(13.20)

# **13.9** Index and Dispersion Offsets

Offsets on refractive index and dispersion may be applied to predefined catalogue materials and fictitious materials. They are entered by the DNO and DVO commands:

DNO delta_ind	Index of refraction offset.
DVO delta_nue	Dispersion offset. The value delta_nue refers to the Abbe-number
	$\nu_d$ (also called V-number) given in absolute values. Example: The $\nu_d$
	value of Schott BK7 is 64.17. A dispersion offset DVO 3.0 results
	in a new dispersion $\nu_d = 67.17$ . For special materials (e.g. infrared
	materials), the actual synthetic $\nu$ -value should be considered when
	specifying DVO. See also the options on fictitious glass models below.
	Defines the model for calculating dispersion offsets used by the DVO
	command. Examples:
	DVOM 1 : Dispersion offsets are exactly calculated according to the
511014 1 4 0	Abbe normal line as defined in the partial dispersion glass diagram
DVOM 1 2	(see sect. 24.3, or command NFNC). Anomalous dispersion of glasses,
	if present, are ignored.
	DVOM 2 : Anomalous dispersion characteristics of special glasses
	is maintained when applying DVO dispersion offsets.

DNO and DVO commands should be applied with great care, since the n and  $\nu$ -offsets are based on standard MIL-glasses (i.e. conform to the so-called ABBE line in the Schott glass diagram). They normally do not take the anomalous dispersion properties of many glasses into account. In addition, DNO and DVO may be used as variables during optimization, to let index and dispersion vary.

Named catalogue glasses that have DNO and DVO offsets assigned are indicated in the surface editor by red colour. In the surface listing (LIS) an asterisk is appended to the glass name. An example is given in Fig. 13.1 and in the listing below.

Standard Data December Tills Apphare GRIN Solves Special Apartures Hologram Mics Array													
orana		Decenter, Tills   A	spri		ves	Special Aperture	2	Hologiani į iš	ansi	c.   Anay			
	TYPE	Radius		Distance		GLASS		APE-Y	×	Shape	GIb	THB	1
OBJ	S	0.0000000		0.1000000E+21				0.00	0	circular	0	0.00000	1
STO	S	131.159656	۷	5.000000		BK7		15.03	0	circular	0	0.00000	Ĩ.
2	S	-150.801750	۷	1.531507				14.94	0	circular	0	0.00000	Ī
3	S	-134.009137	۷	3.000000		SF6		14.80	0	circular	0	0.00000	Ī
4	S	-254.134006	۷	213.0849				14.80	0	circular	0	0.00000	Ī.
IMG	S	0.0000000		·0.3305800E·01	٧			5.26	0	circular	0	0.00000	

Figure 13.1: Glasses with DNO, DVO offsets are indicated by red colour.

#	TYPE	RADIUS	DISTANCE	GLASS		INDEX	APE-Y	AP	CP	DP	ΤP	MP	GLB
OBJ	S	Infinity	0.10000E+21		1.	000000	0.00	С	0	0	0	0	0
STO>	>S	131.1597	5.00000	BK7*	1.	520304	15.03	С	0	0	0	0	0
2	S	-150.8018	1.53151		1.	000000	14.94	С	0	0	0	0	0
3	S	-134.0091	3.00000	SF6	1.	812665	14.80	С	0	0	0	0	0
4	S	-254.1340	213.03629		1.	000000	14.80	С	0	0	0	0	0
IMG	S	Infinity			1.	000000	5.26	С	0	0	0	0	0
GLAS	SS OFFSET	s:											
		DNO	DVO		PGO		PCO		1	4ΙL-	-Cod	de	
#	Index	-offset	Nue-offset	P(g,F)-o:	ffset	P(C,s)−o	ffset						
1	0.00	1500000 -	-2.347000000	0.0000	00000	0.0000	00000		1	5183	3.61	L81	

# 13.10 Partial Dispersion Offsets

Partial dispersion offsets allow the simulation of anomalous dispersion properties of a real or fictitious glass. Since the values to be entered are offsets, PGO and PCO refer to

- the actual partial dispersions in case of a real glass (i.e. a glass from the catalogue)
- the Abbe normal line in case of a fictitious glass.

It should be noted that the partial dispersion offsets are not applicable to gradient index (GRIN) glasses.

#### Command syntax:

PGO delta_P(g,F)	Offset of partial dispersion $P_{(g,F)}$ from the nominal (catalogue) value, in case of fictitious glasses, from the Abbe normal line.
PCO delta_P(C,s)	Offset of partial dispersion $P_{(C,s)}$ from the nominal (catalogue) value, in case of fictitious glasses, from the Abbe normal line.

# 14

# **Image Evaluation**

# 14.1 Geometrical Analysis

## 14.1.1 Paraxial Analysis

A standard collection of paraxial quantities is given in the prescription listing (see LIS command, page 179). These quantities refer to the entire system as indicated in Fig. 14.1. In addition, paraxial quantities may be obtained by specifying surface ranges (si..j) or zoom ranges (zi..j), as described in the table below.

FIR EFL [sij   wij   zij]	Evaluate first orde tion, etc. Retrieve the equiv zoom positions. W is returned for all	r properties, such as focal length, magnifica- valent focal length for a range of surfaces or <i>l</i> ithout parameters, the EFL of the entire system surfaces (s1i), at the reference wavelength,
	for all zoom positi	ons.
	Examples:	
	EFL	! Focal length at reference wavelength, all
		zoom positions
	EFL zl	! Focal length at reference wavelength,
		zoom position 1
	EFL s14	! Focal length of surfaces 1-4, zoom posi-
	z2 w3	tion 2, wavelength 3.
BFL [wk wij zij]	Back focal length	(distance from last surface to image plane)
	at used conjugate	e. Options are for wavelength numbers i to
	j and zoom positi	ons i to j. If a wavelength qualifier (wk) is
	omitted, BFL is re	turned at the reference wavelength.
SEP [zij]	Evaluates the locat	tion of entrance pupil referred to first surface
	(not yet implemen	ted)
SAP [zij]	Evaluates the locat	tion of exit pupil referred to last surface. Op-
	tional at zoom pos	itions zij
		continued on next page

continued from previous page					
SAPI [zij]	Evaluates the reciprocal value of the location of exit pupil, re-				
	ferred to the last surface. That is, $SAPI = 1/SAP$ . This func-				
	tion is particularly useful in optimization where the location of				
	the exit pupil approaches infinity and the SAP function would				
	be discontinuous. Zoom positions zij are optional.				
PRD [zij]	Evaluates the pupil relay distance, that is the axial distance be-				
	tween the entrance and exit pupil. Optional at zoom positions				
	zij				
PRDI [zij]	Evaluates the reciprocal of the pupil relay distance, that is				
	PRDI = 1/PRD. This function is particularly useful in op-				
	timization where the distance between entrance and exit pupil				
	approaches infinity and the PRD function would be discontin-				
	uous.				
OAL sij zij	Overall length: Center thickness between surfaces sij at				
	zoom positions z1				
	setting for OAL is first surface to image for infinite objects, re-				
	Spectively object to image plane distance for limite objects.				
	the first surface in the system				
CVI ci i	Evaluate system length (- sum of thicknesses) for surface range				
	si i If no surface range is specified first surface to last				
	surface (excluding object and image) will be assumed				
OID [sii]	Axial distance from object surface to image surface. If a sur-				
	face range ( $si$ , $i$ ) is specified, the axial distance between sur-				
	faces si j is calculated. For objects at infinity, first surface				
	to image surface is assumed. Note: The previously used com-				
	mand OOS is obsolete but retained for backwards compatibility.				
SH1 [sij] [zij]					
	Evaluates the location of the first (front) principal plane with				
	respect to the first surface specified by s1]. If s1] is				
	lated				
	Evaluates the location of the second (rear) principal plane with				
	respect to the last surface specified by sij. If sij is				
	omitted, the second (rear) principal plane of the entire system				
	is calculated.				
	Related Commands				
UMY sij zij	Paraxial direction angle of the marginal aperture ray (see page				
	108).				
HMY sij zij	Paraxial height of the marginal aperture ray (see page 108).				
UCY sij zij	Paraxial direction angle of the chief ray. See page 108.				
HCY sij zij	Paraxial height of the chief ray. See page 108.				

## 14.1.2 Single Ray Tracing

Tracing a single ray through a system is accomplished by the following commands: sin [ si..j | gk | wi..j | zi..j | fi..j ] ape\_absX ape\_absY



Figure 14.1: Definition of system data

or

rsi [ si..j | gk | wi..j | zi..j | fi..j ] ape\_relX ape\_relY

'sin' traces a single ray given absolute coordinates in the system entrance pupil, whereas 'rsi' traces a single ray based on relative coordinates in the system entrance pupil.

The optional parameter are the designated zoom positions, wavelength, field, surface range and aperture. The ray coordinates at each surface are relative to the local coordinate system of each surface (i.e. the surface vertex).

Specifying a global reference surface gk outputs the ray coordinates with respect to the coordinate system at gk. If global coordinates (see GLO command on page 183) are activated, the ray coordinates are relative to the coordinate system of the surface specified by the GLO-command.

#### Notes on global coordinates output:

The GLO sk command is a permanent command. Once GLO sk is specified, ALL ray coordinates are referred to surface sk any time. Specify GLO N to disable global coordinates output. In contrast, in rsi gk commands (or sin gk commands), global output is active only for this particular command, irrespectively of GLO Y |N| sk settings.

Pupil coordinate definitions:

ape_relX	X-entrance pupil coordinate, a fraction of pupil X-radius. Values are between -1 and +1
ape_relY	Y-entrance pupil coordinate, a fraction of pupil Y-radius. Values are between -1 and +1
ape_absX	X-entrance pupil coordinate, absolute pupil coordinate. Values are absolute in mm.
ape_absY	Y-entrance pupil coordinate, absolute pupil coordinate. Values are absolute in mm.

#### **Examples:**

rsi	f1	w1	g3 0	1	rim ray at field 1, wavelength 1, global ray coordinates re-
					ferred to surface 3
rsi	f1	w1	0 1		rim ray at field 1, wavelength 1, ray coordinates referred to
					local surface coordinates
sin	f1	w1	0 15		rim ray at absolute entrance pupil coordinates $(X/Y = 0/15)$
					at field 1, wavelength 1, ray coordinates referred to local
					surface coordinates

#### 14.1.3 Ray Aiming

aim si [ wi..j | zi..j | fi..j ] ape\_relX ape\_relY

Aims a ray to a specific (relative) aperture coordinate at a given surface si and at the designated zoom positions, wavelengths, and fields. The ray coordinates at each surface are relative to each surface's local coordinate system. If global coordinates (see GLO command on page 183) are activated, the ray coordinates are relative to the coordinate system of the surface specified by the GLO-command.

#### 14.1.4 Single Ray Longitudinal Aberration

LAX [ wij   zij   fij ] ape_relX ape_relY	Computes the longitudinal aberration in the X- plane (sagittal) for a single ray. The aberration is always referred to the image surface.
LAY [ wij   zij   fij ] ape_relX ape_relY	Computes the longitudinal aberration in the Y- plane /tangential) for a single ray. The aberration is always referred to the image surface.

#### Note:

The longitudinal aberration is defined 'along' the optical axis. For ape\_relX = 0 and ape\_relY = 0, i.e. a ray going through the center of the aperture, LAX and LAY correspond to the sagittal and tangential astigmatism for the given fields and wavelengths.

#### 14.1.5 Fan Aberration Curves (RIM Rays)

Fan rays are traced in either tangential or sagittal direction across the pupil. The aberrations may be plotted as transverse or longitudinal aberrations or as optical path difference.

FAN [scale   ?]	Transverse ray aberration fan. The optional parameter
	"scale" sets the aberration scaling for plotting. If not pro-
	vided, the previous scaling value will be used. "?" invokes a
	dialog box to enter the plot scale.
RIM [scale   ?]	as above, only implemented as compatibility mode with CODE
	V.
FANL [scale   ?]	Longitudinal ray aberration fan. The optional parameter
	"scale" sets the aberration scaling for plotting. If not pro-
	vided, the previous scaling value will be used. "?" invokes a
	dialog box to enter the plot scale.
	continued on next page

continued from previous page	
OPDFAN [scale   ? ]	Optical Path Difference (OPD). The aberrations are given in
	fractions of the reference wavelength (wave units). The op-
	tional parameter "scale" sets the aberration scaling for plot-
	ting. If not provided, the previous scaling value will be used.
	"?" invokes a dialog box to enter the plot scale.

The aperture axis in fan aberration plots, i.e. the axis representing the relative aperture coordinates, may be either plotted horizontal or vertical, depending on a users preference. This behaviour can be set in the program preferences (see page 3.2) by selecting from the main menu *File* --> *Preferences* and then checking/unchecking 'Align ray fan curves horizontally' in the operations tab.

## 14.1.6 Spot Diagrams

A spot diagram collects the transverse aberrations in the image plane resulting from tracing a rectangular grid of rays (emerging from a single object point) through the system. Diffraction is ignored. The number of rays traced is approximately proportional to the square of the size of the rectangular grid in the entrance pupil as defined by the NRD command (see page 52). Increasing NRD will increase the accuracy of the spots but will also increase the computation time.

Spot diagrams may be displayed as a function of field, wavelength or zoom position. Note the optional parameter "?", which invokes a dialog box to modify the plot scale, i.e. the scale in which the aberrations are displayed. Alternatively, the plot scale may be specified explicitly as an additional parameter, which is useful in macro sequences.

SPO [plot_scale]	Spot diagram vs. field. This is the default.
SPO LAM [?]	Spot diagram vs. wavelength (colour)
[plot_scale]	
SPO THF [?]	Through Focus Spot diagram. plot_scale is the size
[plot_scale] [def_range]	of the aberration box in the plot and def_range is the
	$\pm$ defocus range along the optical axis.
SPO RIS [?]	Plots ray intersection points on a surface. See also sec-
[plot_scale]	tion 14.1.8.
SPO ZOO [?]	Spot diagram vs. zoom position
[plot_scale]	
SPO FF [?]   [plot_scale] [num_fields]	Array of spot diagrams extending over the full field, where plot_scale is the aberration scale of the spots, num_fields is the number of field points in X-and Y- direction (default = 3) Example: spo ff 0.02 5 ! Plots a 5x5 array of spots, scale is 0.02mm
SPR [fij, wij, zij] SPD [fij, wij, zij]	Evaluates rms-spot radius (SPR) respectively rms-spot diameter at fields fij, wavelengths wij and zoom positions zij. Results are given numerically.

continued from previous page	
SPR FLD [plot_scale ]   [?]	Plots rms-spot diameter versus field. In case of zoomed systems, the currently selected zoom position (see POS command) is used. The maximum of the field definition is used. The question mark "?" invokes a dialog box for entering plot scale, settings of X-or Y-field and reference to chief ray or spot gravity center.
SPR LAM plot_scale [fij]	Plots rms-spot diameter versus wavelength (LAM holds for $\lambda$ ) at fields fij. In case of zoomed systems, the currently selected zoom position (see POS command) is used. The wavelength range is defined by the min- imum and maximum wavelengths used (see WL com- mand). The question mark "?" allows setting of X-or Y-field and reference to chief ray or spot gravity center. <b>Implemented in future release!</b>
SPO [fij   wij   zij] FILE file_name	Write spot aberrations to an ASCII file. No graphic output is generated. The qualifier 'FILE' is mandatory. If file_name is omitted, the user will be asked for a file name. Note that there is no default extension for the file name. The spot aberrations are written in a fixed format with the following columns: pos field colour X-abe Y-abe where pos = zoom position number (integer), field = field number (integer), colour = wavelength number (integer), X-abe = X-aberration relative to chief ray, Y-abe = Y-aberration relative to chief ray.
SPMS marker_size	Temporarily adjusts the size of markers used in spot di- agrams. Marker size is defined in plot units (in mm) re- ferred to the size of a standard A4 paper. The default spot marker size is 0.5mm. The spot marker size is predefined in the preferences section, miscellaneous tab.
IFO incr_in_focus	Increment in focus position

# 14.1.7 Spot Gravity Center

This option calculates the gravity center of the geometrical spot for all fields and wavelengths defined in the optical system.

#### **Example command:**

ygr f3

gives the following output in the "Text Window":

Field	Wavel.	Rel.Wgt	X-Grav.	Y-Grav.	rel.Grav-X	rel.Grav-Y
3	0.54600	1.00	0.00000	18.147916	0.00000	-0.002189
3	0.45000	1.00	0.00000	18.141295	0.00000	-0.008810
3	0.65000	1.00	0.00000	18.146546	0.00000	-0.003559
Weight	ed gravity	center:	0.00000	18.145252	0.00000	-0.004853

The "X-Grav." and "Y-Grav" columns are the absolute gravity coordinates on the image surface referred to the vertex of the image surface. The "rel.Grav-X" and "rel.Grav-Y" columns are the gravity centers referred to the chief ray coordinate at the reference wavelength.

## 14.1.8 Surface Ray Intersection Plot

A square grid of rays, evenly spaced in the entrance pupil, is traced through the optical system and the intersection points of all rays on a designated surface are plotted. See Fig. 14.2. All fields, wavelengths and zoom positions are represented. Rays that are vignetted are not drawn, independently on which surface vignetting occurs. This way, usage of the light beam on a designated surface is shown. The number of rays in the grid are defined by the NRD command. The ray intersection plot is functionally equivalent with the footprint analysis (see page 421), both indicate the area on surfaces used by the beams. Ray intersection plots are more general, because they also take obscurations into account. Due to the finite sampling spacing of the rays, however, the exact boundary of the beam cannot be determined. If precise beam boundaries are required, the footprint option should be used.

SPO RIS [ sk   plot_extent	Plots the intersection points of rays on surface sk. If
? ]	sk is not specified, the default (surface 1) is used on
	the first plot, respectively for subsequent (repeated) plots
	the previously specified surface is used. The parame-
	ter plot_extent is optional and defines the maximum
	displayed area. Absence of plot_extent or a zero
	value invokes automatic determination of the plot extent
	on sk, except where the plot extent has already been de-
	termined by a previous plot. Rays are traced only in the
	reference wavelength.

## 14.1.9 Pupil Intensity Map

The pupil intensity map computes the intensity distribution in the system exit pupil for a given field, wavelength and zoom position. Typically, the intensity distribution across the exit pupil is uniform, however, effects like bulk material absorption or reflection losses at optical surfaces cause a spatial variation of the light intensity in the pupil. In this context, notice that any non-uniform illumination of the system pupil may be considered as *apodization*. Other influences leading to this effect are intensity filters (see INT command, page 140) on surfaces (loaded from an interferogram file, or non-uniform characteristics of the sources itself. For example, laser beams typically exhibit a Gaussian intensity profile which also modifies the effective intensity distribution in the pupil of a system. Summarizing, the pupil intensity plot includes the effects of



Figure 14.2: Ray intersection plot, indicating the area used on a surface. Here shown for a single field.

- Pupil apodization (as defined in system configuration dialog or by PUI command, see page 53),
- Polarization or transmission (see POL and TRA commands, pages ?? and 335),
- Intensity filters, see INT format,
- Coatings and non-uniform coating thickness variations (see CTV).

Plots of the pupil intensity are used to control the intensity distribution in the exit pupil. This is an important feature, as any variation of the system transmission will result in a modification of the image performance. For example, the point spread function (PSF) of most optical systems can be computed by the Fourier Transform of phase and amplitude (the complex field) in the pupil. It is evident that any amplitude modulation will change the form of the PSF.

Pupil intensity maps are obtained by tracing bundles of rays through the entire system and monitor the reduction of the intensity of each ray caused by the above mentioned effects.

Pupil intensity plots are created by the command:

PMA zk fk wk	Pupil map. Plots the intensity distribution across the sys-
[WIR GRY FAL CON XY ?]	tem pupil at field number fk, wavelength number wk
	and zoom position zk. Plots can be displayed as wire
	grid (WIR) which is the default, gray level (GRY), false
	colour (FAL), contour plot (CON) or XY-slices (XY).

The command "PMA ?" (without the quotes) invokes a dialog box for editing plot parameters:

One single plot can be generated for a specific set of field, wavelength and zoom position. The check boxes "*include transmission*" and "*include polarization*" allow overriding of the configuration settings for a particular plot only. For example, unchecking the "*include transmission*" option ignores transmission effects in the pupil map plot, even though transmission analysis (see TRA yes—no command) has been specified. In other words, the settings in this dialog box are temporarily and have no effect on the configuration settings (conditions of use).

The following figures (14.4 to 14.6) show various representations of pupil map intensity.

📢 Pupil Map
Plots the intensity map in the system exit pupil. Transmission and polarization settings are only active for this calculation and do not alter general settings in the system configuration.
Zoom Pos. 1 Show as: Field No. 1 Wire grid Vire grid
☐ Include Transmission ✓ Normalize output plot ☐ Include Polarization
Help Cancel OK

Figure 14.3: Dialog box for editing pupil intensity plot parameters.

#### 14.1.10 Distortion

The distortion is expressed as the coordinate of the real image related to the paraxial image coordinate. It is given in % and may be analysed as chief ray distortion or spot gravity distortion.

$$D = \frac{y_{chief\_ray} - y_{paraxial}}{y_{paraxial}} \cdot 100 \tag{14.1}$$

$$D = \frac{y_{gravity} - y_{paraxial}}{y_{paraxial}} \cdot 100 \tag{14.2}$$

with

$y_{chief\_ray} =$	image height of the real chief ray
$y_{gravity} =$	image height of spot gravity center
$y_{paraxial} =$	paraxial image height (the expected distortion-free image height)

The distortion is always given in %. The paraxial image height  $y_{paraxial}$  is calculated in two different ways:

$$y_{paraxial} = \tan(w) \cdot EFL$$
 for conventional systems, i.e. the image coordinate is propor-  
tional to the tangent of the field angle  
 $y_{paraxial} = w \cdot EFL$  for F-Theta systems, i.e. the field coordinate is proportional to the  
field angle (in radians). This definition is widely used in scanning  
systems.

Afocal systems (i.e. object and image are at infinity) are not adequately described by the equations above. It is more appropriate to define an angular distortion which is the angular deviation of the outgoing beam from a nominal (distortion free) angle. Angular distortion is defined as

$$D_{\alpha} = \frac{\alpha_{real} - \alpha_{paraxial}}{\alpha_{paraxial}} \cdot 100 \tag{14.3}$$

with  $\alpha$  = angle to the optical axis.



Figure 14.4: Pupil intensity map shown in wire-grid (WIR) and gray-scale (GRY) representations. Left: Wire grid plot, command: PMA z1 f2 w3 WIR, Right: Gray scale plot, command: PMA z1 f2 w3 GRY

The so-called F-Theta distortion is only meaningful in systems with an object at infinity. Here, the image height is proportional to the field angle which is mostly required in scanning systems. Strictly speaking, distortion is only valid for centered, rotationally symmetric systems with plane image surfaces, since the paraxial approximation does not account for such special systems.

Vignetting factors are ignored for chief ray distortion. However, for spot gravity distortion, vignetting is taken into account and may have impact on distortion.

Numerical Distortion Analysis		
	Distortion analysis for fie	lds and zoom positions in X-direction.
	The optional parameter	GRAV outputs distortion referred to the
	spot gravity center.	
	Examples:	
DISX [fij, zij,	DISX f13	computes X-distortion at fields 1
GRAV]		to 3
	DISX GRAV f3 w2	computes spot gravity distortion
		in X-direction at field 3 and
		wavelength 2.
DISY [fij, zij,	Distortion analysis in Y-o	lirection.
GRAV]		
FDISX [fij, zij,	F-Theta distortion in X-d	lirection.
GRAV]		
FDISY [fij, zij,	F-Theta distortion in Y-d	irection.
GRAV]		
Distortion Plots		
PLO DISY	Plot distortion in Y-field direction. The entire field extension is	
	plotted.	
PLO DISX	Plot distortion in X-field	direction. The entire field extension is
	plotted.	
		continued on next page

#### **Command syntax:**

continued from previous page	
PLO FDISY	Plot F-theta distortion in Y-field direction. The entire field ex-
	tension is plotted.
PLO FDISX	Plot F-theta distortion in Y-field direction. The entire field ex-
	tension is plotted.
PLO DIG	Plot distortion grid. This is the deformation of a rectangular
	object grid caused by distortion. The full field extension is plot-
	ted. See description below.

## 14.1.11 Grid Distortion Plot :

The distortion grid plot also accounts for non-rotationally symmetric optical systems, which DISX, DISY, FDISX, FDISY do not because they are calculated in the Y/Z-plane only. Calculation of grid distortion assumes a perfectly rectangular grid at the object surface. The distortion of this grid when imaged through the system is then plotted at the image surface (see Fig. 14.7).

This analysis is performed for the full field extension in X- and Y-direction. If only the Y-field is specified (i.e. all X-field coordinates are zero), the full field is assumed circular with the maximum Y-field being the radius of the field circle. A square object field is then inscribed to this circle such that its diagonal (from lower left to upper right corner) is equal to the maximum field circle. The maximum extents of the image are derived from *paraxial* quantities. In extreme wide-angle systems (Fisheye) the paraxial image size may go to infinity if the full field angle approaches 180°, which may lead to problems in the plot diagram. To avoid this problem, a maximum image extension should be provided by the user. The command syntax is

PLO DIG [CHF GRA PSF] [enlargement_factor]	Plots the image of a rectangular object grid. enlargement_factor is the factor by which distortion (i.e. the deviation from the ideal grid) is enlarged in the plot. The distortion grid can be referred to chief rays (CHF), spot gravity centers (GRA) or PSF gravity centers (PSF). The default reference is chief ray (CHF). Examples: plo dig 10.0! plot distortion grid at image sur- face, enlarged by factor 10. plo dig gra 10! as above, however, grid is re- ferred to gravity center of spot.
-----------------------------------------------	--------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------

In particular when distortion is small, the distortion aberration may be enlarged in the plot by a user-defined factor. This may give a better impression of the shape of distortion. The distortion enlargement is defined by

$$x_{plot} = d_f \left( x_{ideal} - x_{real} \right) \tag{14.4}$$

where  $d_f$  is the enlargement\_factor. That is, only distortion aberrations are plotted at an oversized (enlarged) scale, whereas the ideal grid is always plotted at the same size.



Figure 14.5: Pupil intensity maps shown in false-colour (FAL) and contour (CON) representations. Left: False colour plot, command: PMA z1 f2 w3 FAL Right: Contour plot, command: PMA z1 f2 w3 CON

## 14.1.12 Field Aberrations - Astigmatism and Distortion Analysis

The field aberration option computes distortion, astigmatic field curves and optionally longitudinal spherical aberration. It provides a combined plot of all these three types of aberrations. Although longitudinal spherical aberration is not field dependent, it is sometimes desired for traditional reasons.

FIE [LSA] [?]	Plots field dependent aberrations: Astigmatism and distortion.
	The optional parameter LSA also plots longitudinal spherical
	aberration. The question mark invokes a dialog box for set-
	ting aberration scales (enter 0 for automatic scaling). For zoom
	systems the currently selected zoom position is used (see POS
	command). Figure 14.8 shows the plot layout.

Distortion is the change in magnification as a function of field. It is computed from tracing chief rays and is measured in percent relative to the paraxial field height. Astigmatism is represented in terms of longitudinal defocus for tangential (Y) and sagittal (X) planes at various field heights.

In addition to the combined plot, aberrations may also plotted separately. For distortion see sect. 14.1.10, page 247, for longitudinal spherical aberration see sect. 14.1.5, page 242.

## 14.1.13 First Order Analysis

FIR	Lists table of first-order (paraxial) system parameters
	(e.g. EFL, OAL, etc.) for all zoom positions. Note
	that paraxial system data are always output with the LIS
	command. See also the LIS PAR option (page 179).
FIO [sk sij zk zij]	List paraxial data for marginal and chief rays for desig-
	nated surface(s) sk   sij and designated zoom posi-
	tion(s) zk   zij.

Although the ray-tracing equations used in OpTaliX to evaluate an optical system are exact, they are complicated and provide little insight into the image-formation process. To reach simplified analytical results, a *first order* approximation is often a good starting point and in many applications precise enough. This is particularly valid when a common optical axis exists and when the light rays make



Figure 14.6: Pupil intensity maps shown by XY-slices (XY) representations. Command: PMA z1 f2 w3 XY

small angles with the axis. Such rays are called *paraxial rays* and calculations in this domain are denoted as paraxial optics. Paraxial approximations were known already in the early  $17^{th}$  century and Kepler used it when he first formulated the theory of the telescope. Paraxial calculations are derived from Snell's law  $n \cdot sin\theta = n' \cdot sin\theta'$ . If we recall that the sine may be expanded in a series

$$sin\theta = \theta - \frac{\theta^3}{3!} + \frac{\theta^5}{5!} - \frac{\theta^7}{7!} + \cdots$$
 (14.5)

and assuming small values of  $\theta$ , we may approximate  $sin\theta \approx \theta$ . This is the domain of what is called *first-order* or *paraxial* theory.

Paraxial quantities are displayed by the commands LIS, LIS PAR or FIR. For a detailed description of the output values see section 9.1 (page 179).

## 14.1.14 Third Order Analysis (Seidel Aberrations)

Third order aberrations are an approximation to the aberrations obtained by real (skew) ray trace. The advantage of third order<sup>1</sup> aberrations is that they can be calculated easily and quickly on the basis of paraxial quantities. In the contrary, exact ray trace equations are complicated as they involve the trigonometric functions of angles, instead of just the angles. When we speak of third order approximation, we truncate the series expansion given in Eq. 14.5 after the  $\theta^3$  term and only the first and third order terms in the expansion of the sine are retained. The resulting equations and corresponding aberrations are part of *third order optics*. In the same way that the sine was expanded in a series, the aberrations can be expanded. The first term in the expansion is known as the *third order aberration* (i.e. the first approximation to the total aberration).

To illustrate this point, Fig. 14.9 shows the spherical aberration of a lens based on real ray trace data. The aberration curve based on third order equations is shown as thick line.

Fig. 14.9 indicates that third order aberrations only give a more or less coarse approximation to the real aberration, in particular for larger apertures and/or fields. This behaviour depends on the system used. The beauty of third order aberrations, however, must be seen in the fact that they provide a deeper insight into the contributions of each surface onto the overall aberration of an optical system.

The astute reader may argue that an approximation involving fifth order aberrations may simulate the aberrations much better and give an even more deeper insight. However, fifth order (or even 7th order) equations are nearly as complex as real ray trace equations. Due to the advent of fast computers,

<sup>&</sup>lt;sup>1</sup>sometimes also referred to as *tertiary* aberrations


Figure 14.7: Grid distortion plots. Left: Distortion referred to chief rays. Right: Distortion referred to spot gravity center.

exact ray trace aberrations, which include *all* orders, can be computed equally fast and there is no convincing reason any more to using  $5^{th}$  order or higher order aberrations.

#### **Command:**

THOOutputs the third order (Seidel) aberrations with surface contributions.	
-----------------------------------------------------------------------------	--

#### **Third Order Formalism:**

We refer to the paraxial quantities established in section 5.3 and define some system constants:

$$H = nu_a h_b - nu_b h_a \quad \text{(Helmholz-Lagrange invariant)} \tag{14.6}$$

$$S = \frac{Y'}{2H} \tag{14.7}$$

$$S_p = \frac{Y' \cdot \Delta\omega}{H} \tag{14.8}$$

$$S_s = \frac{Y'}{H} \cdot \left(\frac{\Delta\omega}{2}\right)^2 \tag{14.9}$$

The paraxial image height is Y' and the Buchdahl chromatic variable  $\omega$  is defined as (see [7],[46]),

$$\omega = \frac{\lambda - \lambda_0}{1 + 2.5 \left(\lambda - \lambda_0\right)} \tag{14.10}$$

where  $\lambda_0$  is the reference wavelength. For each surface, we define the following auxiliary variables:



Figure 14.8: Field aberrations, astigmatism, distortion and longitudinal spherical aberration, combined in one plot.

$$i = c \cdot h_a + u_a \tag{14.11}$$

$$j = c \cdot h_b + u_b \tag{14.12}$$

$$b_a = \frac{n}{n'} (n - n') h_a (u_a + i)$$
(14.13)

$$b_b = \frac{n}{n'} (n - n') h_b (u_b + j)$$
(14.14)

$$a = (n - n') (k \cdot c^3 + 8A_4)$$
(14.15)

$$d_p = \frac{\partial n}{\partial \omega} - \frac{n}{n'} \cdot \frac{\partial n'}{\partial \omega}$$
(14.16)

$$d_s = \frac{\partial^2 n}{\partial^2 \omega} - \frac{n}{n'} \cdot \frac{\partial^2 n'}{\partial^2 \omega}$$
(14.17)

From these constants, we obtain the surface contributions to the third order (Seidel) aberrations:

spheric terms:

#### aspheric terms:

Spherical: $A_i =$	$S \cdot b_a \cdot i^2$	+	$S \cdot a \cdot {h_a}^4$
Coma: $B_i$ =	$S \cdot b_a \cdot i \cdot j$	+	$S \cdot a \cdot h_a{}^3 \cdot h_b$
Astigmatism: $C_i =$	$S \cdot b_a \cdot j^2$	+	$S \cdot a \cdot {h_a}^2 \cdot {h_b}^2$
Petzval: $P_i =$	$S \cdot H^2 \cdot \frac{n-n'}{n \cdot n'} \cdot c$	+	0
Distortion: $V_i =$	$S \cdot \left[ b_b \cdot i \cdot j + H \left( u_b'^2 - u_b^2 \right) \right]$	+	$S \cdot h_a \cdot h_b{}^3$
Axial Color: $Fl_i =$	$S_p \cdot d_p \cdot h_a \cdot i$	+	0
Lateral Color: $Fq_i =$	$S_p \cdot d_p \cdot h_a \cdot j$	+	0

The third order aberrations of the entire system are then the sum of the corresponding aberration contributions associated with the individual surfaces of the system, hence



Figure 14.9: Third order aberration in comparison to real ray trace data, shown on the example of spherical aberration.

$$SPA = \sum_{i=1}^{n} A_i \tag{14.18}$$

$$COMA = \sum_{i=1}^{n} B_i \tag{14.19}$$

$$ASTI = \sum_{i=1}^{n} C_i \tag{14.20}$$

$$PETZ = \sum_{i=1}^{n} P_i \tag{14.21}$$

$$DIST = \sum_{i=1}^{n} V_i \tag{14.22}$$

$$LCA = \sum_{i=1}^{n} Fl_i \tag{14.23}$$

$$TCA = \sum_{i=1}^{n} Fq_i \tag{14.24}$$

## 14.1.15 Secondary Spectrum

The secondary spectrum (longitudinal colour) is the variation of the *paraxial* focus along the optical axis as a function of wavelength.

SSP	Secondary Spectrum, numerical output. Since this analysis is
	based on paraxial calculations, results may not be meaningful
	for non-paraxial (tilted, decentered or off-axis) systems.
PLO SSP [ plot_scale	Plots the secondary spectrum. The optional question mark "?"
? ]	invokes a dialog box for entering the plot scale.
SSR [wij   zij]	Secondary spectrum, weighted rms-value. It is computed as the
	rms-variation of the paraxial focus at wavelengths wij (in-
	cluding spectral weights) and at zoom positions zij. Since
	this analysis is based on paraxial calculations, results may not
	be meaningful for non-paraxial (tilted, decentered or off-axis)
	systems.

For a given wavelength, the lateral colour is the distance on the image surface with respect to the reference wavelength. A curve is plotted for each wavelength. Chief rays are used for this analysis.

Quite often the lateral colour is defined as the distance on the image surface from the shortest wavelength to the longest wavelength chief ray intercept. However, a lot of information is lossed by this approach, which may be misleading because the shortest/longest wavelength may not exhibit the worst aberration. This problem is avoided in OpTaliX.

LAC wij [fij,	Lateral colour within wavelength range wij. A wavelength
zij]	range is required, field and zoom specification are optional.
	It is the maximum lateral deviation for all wavelengths from
	the chief ray intercept of the ray at the reference wavelength.
	Wavelength weights are not in effect for this type of analysis.
PLO LAC	Plot lateral colour vs. field. For each wavelength, the lateral
	deviation from the chief ray intercept of the ray at the reference
	wavelength is plotted vs. field. A dialog box is opened to enter
	the plot scale.

## 14.1.17 Ghost Image Analysis

Optical systems can form unintended images due to reflections between pairs of surfaces. All lens surfaces reflect light to an extent depending on the refractive index of the glass itself respectively on the type of anti-reflection coating applied to these surfaces. Light reflected from the inner surfaces of a lens will be reflected again and may form reasonably well-defined images close to the image surface. Such spurious images are called *ghost images*.

The number of possible surface combinations (pairs) which may contribute to ghost images is n(n-1)/2, where n is the number of lens surfaces in the system. As the number of surfaces grows, the probability of ghost problems also increases. For example, a zoom lens with 10 lenses (20 surfaces) gives 190 possible ghost images.

As a guideline, the transmittance of a lens including all possible multiple reflections, but ignoring any loss of light by absorption in the glass, is given by [22]

$$t = \frac{1 - r}{1 + (N - 1)r} \tag{14.26}$$

where r is the reflectance of each surface and N is the number of surfaces. Thus, the reflected portion (1 - t) does not contribute to the image formation, it is considered stray light. On the example of the above mentioned zoom lens with 20 air-glass interfaces, the amount of ghost radiation compared to the total radiation passing the lens is 45% for uncoated surfaces and about 17% if the surfaces are anti-reflection coated (1% reflection loss).

Most of this ghost radiation is harmless if it is diffuse enough, i.e. spread uniformly over the entire image area. However, if brought to focus near the image surface, ghost images can be quite intense even in case of anti-reflection (AR) coatings. It is therefore of utmost importance to control not only the amount of ghost (stray) radiation but also its intensity distribution.

OpTaliX provides four types of analyses to study the effects of ghost images.

• Paraxial Analysis: Find the *paraxial* location and apparent diameter of the ghost image with respect to a target surface (typically the image surface, but can be any other surface as well).

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- Calculate the spot diagrams based on exact ray trace along the ghost path (including the internal double-reflection).
- Plot a lens layout showing the ghost path.
- Create a photo-realistic image of ghost effects, including effects of anti-reflection coatings and ghost spot distribution.

GHO SUR sij	Ghost surface range. The surfaces sij denote the
	first and last surface to be included in ghost analysis.
GHO TAR sk [x_ext, y_ext]	Target surface at which ghost effects are to be ana-
	lyzed. The optional parameter x_ext, y_ext define
	the extension of the analysis area at the target sur-
	face.
GHO SRC	Include the effects of the source. That is, the analysis
	includes the irradiation at the target surface caused
	by the source itself <b>plus</b> the effects caused by ghost
	radiation. Since the expected intensity differences
	between direct image and ghost image may be large,
	logarithmic display is recommended (see GHO LOG
	command below).
GHO LOG [Y N]	Logarithmic display of ghost intensity. Y enables
	logarithmic display, N disables it (i.e. resorts to lin-
	ear scale). Note the GHO FLOOR command below.
	Defines the lowest intensity level $I_{min}$ that
	can be displayed in logarithmic display (re-
	quires GHO LOG Y). $I_{min}$ can be specified
	as linear or logarithmic value: Negative num-
	bers are considered as $log(I_{min})$ , positive
GHO FLOOR i_min	numbers as linear value.
	Examples:
	gho floor -3 ! Lowest relative intensity
	is $10^{-3} = 0.001$ ,
	gho floor 0.001 ! Lowest relative in-
	tensity is 0.001
GHP sij target_sur [ALL]	
GHO sij target_sur [ALL]	Find the <i>paraxial</i> location and apparent diameter
	of the ghost image with respect to a target surface.
	sij are the first and last surface where ghost re-
	flections take place. The optional parameter ALL
	lists all possible surface pairs within the surface
	range sij. The commands GHP and GHO are
	functionally equivalent. GHO was added for compat-
	ibility with Code V. See also the notes on paraxial
	ghosts below.
	continued on next page

continued from previous page	
GHS sij target_surf GHO SPO sij target_surf	Calculate the spot diagrams based on exact ray trace along the ghost path. sij are the first and last surface where ghost reflections take place. The target surface target_surf may be any surface includ- ing the image surface.
GHV sij target_surf GHO VIE sij target_surf	View lens layout plot including ghost ray trace. sij are the first and last surface where ghost re- flections take place.
GHR sij target_surf x_rel_aperture y_rel_aperture GHO RAY sij target_surf x_rel_aperture y_rel_aperture	Trace a single ghost ray. sij are the first and last surface where ghost reflections take place.
GHO RGB sij target_surf [ALL] [FILE file_spec]	<ul> <li>Calculate an almost photo-realistic RGB-image. sij are the first and last surface where ghost reflections take place. The optional parameter ALL includes the ghost contributions of all possible surface pairs within the surface range sij, including coating effects (requires POL Y), transmission effects (requires TRA Y) and the spectral weighting of the system.</li> <li>The optional parameters FILE file_spec allow export of the ghost RGB data to a file specified in file_spec. Two formats currently supported are plain ASCII and Microsoft<sup>TM</sup> Excel. The file format is derived from the file extension, i.e. a file name test.xls will create an Excel file, whereas any other extension defaults to ASCII.</li> <li>More information about "photo-realistic rendering of ghost effects" is also given on page 259.</li> <li><b>Example:</b> gho rgb s37 12 all fil c:\temp\ghostrgb.xls</li> </ul>
GHO SAV Y N	Save ghost analysis parameters along with optical system prescription.

## Limitations:

The current implementation of ghost analysis (respectively the underlying inverse ray trace) takes spherical surfaces, aspheric surfaces and decentered and/or tilted surfaces into account. Gradient Index (GRIN) media are also correctly simulated in the inverse ray trace, however, the end surfaces of GRIN elements must be centered.

## 14.1.17.1 Notes on paraxial ghost analysis:

Ghost analysis based on paraxial calculation provides a very fast means for identifying the most disturbing surface pairs. However, the results of paraxial ghost analysis should be observed with great care, because paraxial analysis does not account for geometrical aberrations along the ghost path. Ghost images, however, are not corrected to produce sharp images. Therefore, the more common case is that ghost images are blurred by large amounts of spherical aberration, coma and field curvature.

It is therefore likely that the effect of ghost images predicted by *paraxial* analysis does not match well with an exact ghost ray trace. Only for optical systems that exhibit small numerical apertures and small fields only, paraxial ghost quantities may reasonably represent real ghost effects. As an example, the paraxial ghost analysis shown below exhibits a relatively small ghost spot for the surface pair 5-7 (that is, first reflection is on surface 7, second reflection is on surface 5). However, the exact ghost ray trace, as shown in Fig. 14.10, reveals a large spread of the rays on the image surface caused by severe (uncorrected) spherical aberration along the ghost path.

Note that the often observed discrepancy between paraxial ghosts and *real* ray trace ghosts is not an implementation fault in OpTaliX but is *only* due to the inherent limitations of paraxial theory (i.e. linear approximation of real world effects).

Thus, be warned NOT to trust paraxial ghost analysis as the sole means of performing ghost analysis, because it is fast, but always cross-check results of paraxial ghost analysis against other methods (for example ghost spot, ghost lens view or ghost RGB-analysis).

PARAXIAL GHOST ANALYSIS:



Figure 14.10: Ghost imaging. Note the spread of the rays on the image surface due to (uncorrected) spherical aberration along the ghost path as opposed to the size of the ghost image predicted by paraxial analysis.

Thus, the user should be aware of the intrinsic limitations of paraxial ghost analysis, which may be appropriate in "slow" systems but may fail in systems with large numerical aperture or systems having a wide field.

### **Example:**

The following example uses a Double-Gauss system (see *\$i\examples\misc\double\_gauss-2.otx*). First reflection takes place on surface 7, directing the rays backwards. The second reflection takes

place on surface 5, directing the ghost rays back to the image surface. The ghost ray trace is visualized by the command

ghv s5..7 12

where s5..7 defines the surface range. The third parameter is the target surface (12). Fig. 14.11 shows the nominal imaging ray trace and the corresponding ghost ray trace for the surface pair 5 and 7. Also note the surface numbers, which are identical for both cases, indicating that extra surfaces (which describe the ghost path) are not required.



Figure 14.11: Ghost imaging. Left: conventional imaging path, right: ghost imaging path between surfaces 5 and 7.

#### 14.1.17.2 Photo-realistic rendering of Ghost Effects:

The "GHO RGB" option provides the most realistic and accurate ghost analysis. It offers a fully automatic search of ghost effects by evaluating *ALL* possible combinations of surface pairs in a lens which may contribute to ghosts. If enabled, the analysis also includes wavelength dependent effects of multi-layer coatings on optical surfaces ("POL yes"), material absorption ("TRA yes") and vignetting.

The colors in the RGB-plot are approximate to the 'real world' colour rendition only for systems in the visible spectral range, that is approximately 400 - 700 nm. If other spectral ranges are used (for example ultra-violet or infrared spectral regions), then a 'blue' colour in the plot only represents a shorter wavelength in that spectral range, respectively a 'red' colour corresponds to a longer wavelength. In such cases, colors should be considered as 'pseudo' colors only.

In order to create photo-realistic plots of ghosts, some preparatory work is recommended:

- We define a single object which is considered as the disturbing source, being either inside the specified field of view or outside.
- All surface apertures should be fixed (FHY sa 1) so that ghost rays hitting a surfaces outside its defined aperture are effectively blocked.
- Coatings should be appropriately attached to surfaces (see ATT command) in order to model ghost reflections realistically.
- Polarization and transmission analysis must be enabled (POL Y, respectively TRA Y) to include effects of coatings in the ghost analysis. POL and TRA may also be set separately in the



Figure 14.12: Almost photo-realistic rendering of ghost effects as a RGB-image on the example of \$i\examples\high\_na\f15\_33.otx. The left image was obtained by ignoring coating or Fresnel reflection effects, whereas the right image is more realistic by including coating effects (POL Y, TRA Y)

ghost analysis dialog. Note that polarization calculation is computationally intensive, which may slow down the speed of the calculation by an order of magnitude. Therefore, it is sometimes helpful to do a first ghost analysis with POL and TRA disabled and study the geometrical effects of ghosts only. For a detailed and precise analysis, POL and TRA should be enabled to include the intensities of ghost images. For the differences of enabled/disabled coatings see Fig. 14.12.

For each pair of ghost surfaces the RGB-ghost analysis outputs the location and the relative intensity of the ghost image. This information helps to identify contributions to the ghost image from particular surface combinations. A typical output from a RGB-ghost analysis would be:

Surface se	equence:	0> 4>	3> 21	
WL	Rays	X-grav.	Y-grav.	Rel.Int.
0.55000	) 187	2.59402	2.19795	0.00000506
0.43000	) 186	2.66335	2.25453	0.000003985
0.62000	) 187	2.58922	2.19467	0.00000319
Surface se	equence:	0> 5>	1> 21	
WL	Rays	X-grav.	Y-grav.	Rel.Int.
0.55000	) 97	2.25870	2.26849	0.00000940
0.43000	) 95	2.26453	2.25057	0.000001150
0.62000	) 97	2.26605	2.27590	0.00000163
Surface se	equence:	0> 5>	2> 21	
WL	Rays	X-grav.	Y-grav.	Rel.Int.
0.55000	) 145	-2.21976	-2.28230	0.000001083
0.43000	) 145	-2.10141	-2.16481	0.00000826
0.62000	) 145	-2.25932	-2.32177	0.00000173

Output is given for each wavelength defined in the system. The "X-grav" and "Y-grav" coordinates are the intensity-weighted gravity centers of the ghost image at the target surface. It helps to easier identify the location of a particular ghost in the RGB-image. The relative intensity (Rel.Int.) column gives the average intensity of a particular ghost in relation tho the intensity of the light entering the optical system. The Rel.Int. column does not give a measure of the ghost irradiance on the target surface.

### 14.1.17.3 Writing Ghost Data to Files (ASCII or Excel

Irradiance distributions resulting from photo-realistic Ghost RGB (red-green-blue) analyses may also be written to a file. The supported file formats are Excel (.XLS), or ASCII (.TXT or .DAT), whereas

the file format is derived from the extension itself.

On export, all channels are written successively into a single file, that is, red, green, blue channels and the composite "white" channel.

#### **ASCII-Format:**

Each channel of the Ghost RGB image is preceded by two comment lines indicating the channel and the maximum ray intensity (max value) in that channel. Data of each channel are then written normalized with respect to the channel maximum intensity. The typical output format is shown below:

```
! red:
! max value = 581.4250488281250
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
! green:
! max value = 406.000000000000
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
! blue:
! \max value = 635.9754028320312
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 0.00000 .....
! white:
! \max value = 1623.400390625000
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
0.00000 0.00000 0.00000 0.00000 0.00000 0.00000 ....
0.00000 0.00000 0.00000 0.00000 0.00000 .....
```

### **Excel-Format:**

Images from ghost RGB analyses may be written to Excel. Each red-green-blue component of the ghost image is then written to a separate sheet in the Excel file. The fourth channel "white" is a composite of the three RGB channels.

## 14.1.18 Vignetting Analysis

Vignetting is a reduction in the size of the entrance pupil, for off-axis fields, because several surfaces may limit the transverse extension of the beam. Using this definition there is no vignetting on-axis.

53	4.311024	11.49606	26.86614	31.17717	11.49606	4.311024	4.748032
54	5.748032	12.93307	57.48032	63.22835	12.93307	5.748032	4.311024
55	5.748032	15.80709	177.189	200.1811	15.80709	5.748032	5.748032
56	8.622047	11.93307	43.11024	48.85827	11.93307	8.622047	5.748032
57	7.18504	11.05906	20.11811	24.42913	11.05906	7.18504	5.748032
58	6.18504	10.05906	7.18504	10.05906	10.05906	6.18504	2.437008
59	5.748032	5.748032	5.748032	8.622047	5.748032	5.748032	1.437008
60	2.874016	5.748032	4.311024	8.622047	5.748032	2.874016	1.437008
61	0	0	2.874016	4.311024	0	0	0
H 4	🔸 🕨 🔪 Tab	elle1 / Tabe	lle2 / Tabell	e3 $\lambda Red / \cdot$	Green / Blue	/ White /	•
Berei	it						

Figure 14.13: The RGB components from ghost images are written to separate tabs in an Excel file, including the composite "white" channel. The preceding tabs labeled "Tabelle1" to "Tabelle3" are dummy sheets and should be ignored.

Vignetting leads to a decrease of the illuminance of the image towards the edge of the field. Also, vignetting is often used in the design stage to have a better control of aberrations.

In OpTaliX vignetting properties of an optical system are *solely* defined by surface apertures which have the "fixed height" property assigned (see FHY command, page 171). Vignetting analysis is always referred to the first field (F1) in the field list, which, for centered systems, is assumed the axial case. For non-centered systems, i.e. systems which contain decentered/tilted surfaces or have a non-symmetrical field, the reference field must be specified in the first position (F1) of the field list.

#### **Commands:**

VIGP	Plots vignetting as a function of field. In case of zoom systems, all vignetting is overlayed for all positions in a single plot.
VIG [fij wij zij]	Evaluate vignetting numerically at discrete fields fij, and zoom positions zij. Vignetting is always integrated and spectrally weighted over wave- lengths wij. Values are returned between 0 (100% vignetting) and 1 (no vignetting). By that definition, it is a measure of relative illumination. If fields are not spec- ified, the maximum field will be used. If zoom positions
	always integrated and spectrally weighted over wave- lengths wij. Values are returned between 0 (100% vignetting) and 1 (no vignetting). By that definition, it is a measure of relative illumination. If fields are not spec- ified, the maximum field will be used. If zoom positions are not specified, zoom position 1 is used.

### 14.1.19 Geometric Modulation Transfer Function

Calculates the geometrical approximation of the modulation transfer function (MTF). This analysis is appropriate when the wavefront aberration is large compared with the wavelength. We may then approximate the optical transfer function (MTF) by [34]

$$\hat{H}(f_x, f_y) = \iint_{-\infty}^{+\infty} A(x, y) e^i (\Delta x \omega_x + \Delta_y \omega_y) dx, dy$$
(14.27)

where

$$\begin{aligned}
\omega_x &= 2\pi f_x \\
\omega_y &= 2\pi f_y
\end{aligned} \tag{14.28}$$

and  $\Delta_x, \Delta_y$  are the transverse aberrations,  $f_x, f_y$  are the spatial frequencies of interest and A(x, y) is the relative amplitude associated to each ray. The geometric aberrations  $(\Delta_x, \Delta_y)$  are obtained from tracing a bundle of rays through the system, rectangularly gridded across the entrance pupil. With this assumption, by dividing the aperture in small squares, the geometrical transfer function may be written as

$$\hat{H}(f_x, f_y) = A(x, y) \left\{ \sum_{i=1}^N \cos(\Delta_x \omega_x + \Delta_y \omega_y) + \sum_{i=1}^N \sin(\Delta_x \omega_x + \Delta_y \omega_y) \right\}$$
(14.29)

where the sum is performed for all rays N on a spot diagram. This geometrical approximation is surprisingly accurate when the aberrations are larger than a few wavelength. In very well corrected systems, for example where geometric aberrations are in the order or smaller than the Airy-diameter, the geometric approximation of the MTF yields better results than are physically possible. The diffraction based MTF should be used instead (see section 14.2.1, page 270).

MTF FRE FLD DEF [NUM] GEO	Geometric MTF. The optional parameters can be spec- ified in any order. Note that polarization effects are ig- nored for geometrical response calculations. Examples: MTF FLD GEO ! geometric MTF vs. field, MTF GEO FLD NUM ! only numeric output of geom. MTF vs. field.
GMTFT [fk zk]	Tangential geometric MTF at field fk, zoom position zk. For use in optimization, UGR and EVAluation commands only.
GMTFS [fk zk]	Sagittal geometric MTF at field fk, zoom position zk. For use in optimization, UGR and EVAluation commands only.
GMTFA [fk zk]	Average geometric MTF at field fk, zoom position zk. GMTFA = 0.5(GMTFT + GMTFS). For use in opti- mization, UGR and EVAluation commands only.

## 14.1.20 Geometric Point Spread Function (GPSF)

The GPSF analysis is a purely geometric approximation to the image of a point source. Since only ray aberrations are included, diffraction effects are completely ignored. This analysis may be useful in systems where aberrations are large compared to the diffraction limited performance. Use the PSF option (page 273) if diffraction effects shall be taken into account.

This analysis includes spectral weighting (as defined in the system configuration), transmission effects (requires POL yes and TRA yes) and aperture apodization.

By default, the calculation is performed for all fields and wavelengths defined in the system configuration.

	Geometric point spread function. This analysis is based on geometric effects only. It is most appropriate where aberrations are large. Use the PSF command (see page 273) to include diffraction effects. img_size is the patch size at the image surface. Plot options:
GPSF zk fij wij img_size [VIE CON FAL XY] [?]	<ul> <li>VIE: perspective plot (wire grid),</li> <li>FAL: "false" colour geometric PSF. The intensity of the PSF is coded into a rgbmodel. Blue colour represents low intensities, red colour represents high intensities.</li> <li>CON: contour plot of geometric PSF</li> <li>XY: cross sectional plots (in X- and Y-direction)</li> </ul>
	GPSF traces grids of rays for all fields and wavelengths specified and plots the <i>relative</i> intensity in the image plane.
GNRD num_rays_diam	Number of rays across diameter for geometric PSF calcula- tions only. Note that GNRD is equivalent to NRD, however, it is effective only during GPSF-calculations. Also, GNRD does not change NRD. Any positive number for GNRD is allowed.

### Example commands:

GPSF	f23 0.05 FAL	Calculates geometric PSF for fields 2-3. Intensity distribution is shown on a 0.05mm image patch as false-colour coded image.
GNRD	30	sets number of rays across diameter for GPSF calculation exclusively.
GPSF	?	invokes a dialog box for adjusting parameters prior to calculating GPSF.

## 14.1.21 Encircled Energy (Geometric)

Calculates the fraction of energy by counting all rays that pass the optical system (i.e. are not vignetted) and hit the image surface within a specified area (defined by its diameter). An evenly-spaced rectangular grid of rays in the entrance pupil (see NRD) is traced to the image surface for specified wavelengths, field and zoom positions. Each ray is assigned an energy proportional to its wavelength weight (WTW), aperture apodization and relative transmission.

RAD fij [wij] diam_x [diam_y] [X posx Y posy]	Fraction of energy contained in an image area defined by diam_x, diam_y. Solely based on geometrical analysis, diffraction is ignored. For diffraction encircled energy see ECE command (page 285). If diam_y is omitted (that is only diam_x is specified), the image area is assumed circular. Both values, diam_x and diam_y must be specified for a rectangular/square area. The center of the image area is assumed to lie at the location of the chief ray coordinates in the im- age plane, except when the optional parameter set [X posx Y posy] is specified (see below). In- cludes wavelength weight (WTW), transmission and apodization.
	The optional parameter set [X posx Y posy] clamps the specified area at a fixed position (posx, posy) on the image surface rather than defining the area with respect to the chief ray locations for each field. This way, rays are integrated on the same area for all fields and zoom positions.
ECG fij zk image_radius [NUM GRV]	Plots geometric encircled energy. Entirely ray based analysis. Takes into account transmission (see TRA/POL) and apodization effects (see PUI/PUX/PUY), if enabled. Use the NUM option to list numerical values. The optional parameter GRV refers analysis to the spot gravity center. If omitted, the chief ray reference at the designated fields, respectively the last setting is used. Two curves are plotted, one for the geometric energy contained in a defined image circle ( <i>encircled</i> energy) and one contained in a defined square ( <i>ensquared</i> energy). See also Fig. 14.14 for the expected plot.

### **Examples:**

RAD f3 0.01 0.02	! Output geometric encircled energy at field 3 contained in a rectangular area of $X = 0.01$ mm, $Y = 0.02$ mm.
eva [RAD f3 0.01 0.02]	! Evaluate geometric encircled energy at field 3 contained in a rectangular area of $X = 0.01$ mm, $Y = 0.02$ mm.
RAD f14 .5 X 0.0 Y 0.0	! Geometric encircled energy within a circular area of
	0.5mm diameter with fixed location at $X = 0$ , $Y = 0$ .
ECG f12 z3 0.1 NUM	! Plot geometric encircled energy at fields 1-2, zoom posi-
	tion 3, image diameter 0.1mm and report numerical values.

## 14.1.22 Quadrant Detector Analysis

The quadrant detector analysis (QUA) option shows the scanned response of a quadrant detector to the image at each field. As in all geometric analyses, diffraction effects are ignored.



Figure 14.14: Encircled Energy geometric (ECG). Plots the fraction of energy associated to rays that hit a defined circle (or square) at the image surface. Includes transmission and apodization effects.

A quadrant detector is a semiconductor photodiode divided into four sensitive areas. Such devices are typically used to provide alignment information, as determined by comparisons of the illumination levels of opposing quadrants.

The computation lists the scanned response of a simulated quadrant detector to the image at each field point. Scanning is done for both X- and Y-directions. It assumes proper coupling of the quadrants in each half. See Fig. 14.15.

QUA [STE scan_step_size] [fij] [zk]	Quadrant detector analysis, showing the scanned response of a quadrant detector to the image at fields fij and zoom position zk. Diffraction is ignored.
QST scan_step_size	Quadrant step size, in lens units at the image plane.
QSM smooth_diam	Gaussian smoothing diameter, in lens units.

### Notes:

Quadrant detector analysis is based on the number of rays across the pupil diameter (NRD) and it takes into account apodization and wavelength weights. If enabled (TRA Y and/or POL Y), transmission and polarization effects are also taken into account.

The scanned response may be smoothed by a small spot of Gaussian shape. The diameter of the smoothing Gaussian (QSM) is defined at an intensity 50% of the peak intensity.

### **Description of Output:**

In addition to the plot output, a listing is generated for each field activated (see FACT command). The listed output shows the response of the two detector halves in X- and Y-direction as well as the ratio



Figure 14.15: Movement of the halves of a quadrant detector across the spot at a given field. Shown are the two scan directions, in X (left) and in Y (right).

of responses from the two halves of the detector as a function of the scan position. As an example, we will restore the "Double-Gauss" file from the examples library (\$i\optalix\examples\double\_gauss.otx). The settings are QST 0.02 and QSM 0.02. Plot and numerical output are invoked by QUA f1.

```
QUADRANT DETECTOR ANALYSIS:
```

Field : 1	X = 0.00	000 Y =	0.00000
X-Shift	Left Half	Right Half	Ratio
-0.06000	0.00000	1.00000	0.00000
-0.04000	0.00250	0.99750	0.002507
-0.02000	0.02293	0.97707	0.023464
0.00000	0.47937	0.52063	0.920737
0.02000	0.97707	0.02293	42.618182
0.04000	0.99750	0.00250	398.833333
0.06000	1.00000	0.00000	1000000.000000
Y-Shift	Left Half	Right Half	Ratio
-0.06000	0.00000	1.00000	0.00000
-0.04000	0.00250	0.99750	0.002507
-0.02000	0.02293	0.97707	0.023464
0.00000	0.47937	0.52063	0.920737
0.02000	0.97707	0.02293	42.618182
0.04000	0.99750	0.00250	398.833333
0.06000	1.00000	0.00000	1000000.000000

## 14.1.23 Biocular Analysis

The term "biocular" relates to viewing viewing with both eyes simultaneously. This term must not be confused with "binocular" systems. In biocular systems, both eyes look through the same optical system, in binocular systems, the human eyes look through two identical (mirror symmetrical) optical systems (telescopes), mounted side-by-side. The latter is often denoted as "Feldstecher" (German) or field glasses.

The biocular analysis (BIO) is useful in optical systems that provide an enlarged image of a display and which is observed from different (typically two) eye locations. The BIO option computes chief rays over a grid of viewing angles and displays the differences of the images. Essentially, a biocular magnifies a small display and presents the enlarged image to the visual system. Biocular systems are viewed through with both eyes simultaneously (as opposed to binocular systems). Other typical applications of the BIO option are head-up-displays (HUD) and simulators.

The BIO option allows analysis of the following parameters:

- Convergence: The human eyes are focusing to an object at a distance closer to infinity, that is the simultaneous inward movement of both eyes toward each other.
- Divergence: The human eyes are focusing to an object in excess of infinity distance (i.e. a virtual image) and the eyes are forced to simultaneously move outward with respect to each other. This is a situation that the eyes cannot perform and that leads to eye strain and headache.
- Dipvergence: The two images observed by the eyes are laterally displaced in vertical directions. Again, this may lead to eye strain and headache.
- Biocular FOV: The angular range within observation of the display is possible with both eyes simultaneously. Typically, the FOV seen by the left or right eyes are different and do only partly overlap. The "biocular FOV" is only the overlapping region.

The locations of the left and right eye are modelled via two zoom positions. The aperture stop is usually at the eye locations in front of the optics and is decentered to model the standard interpupillary eye distance of 64mm. The first zoom position decenters the stop -32mm in X-direction for the left eye while the second zoom position decenters it +32mm in X-direction for the right eye. The stop diameter is set in accordance to the diameter of the eye pupil (typically 5mm). Figure 14.16 indicates the preferred condition.



Figure 14.16: Optical setup for biocular analysis. Left and right eyes are modelled by small decentered apertures via two zoom positions.

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BIO FOV CON DIP [? NUM]	DIP : Plot dipvergence NUM : optional parameter, outputs numerical data. Example: BIO FOV NUM ? : Plots biocular FOV, outputs numerical data and invokes a dialog box for setting analysis parameters
BIO FOVX FOVY fov_min fov_max	Defines field-of-view (FOV) in horizontal (FOVX) or vertical (FOVY) direction. Values must be given in de- grees. Examples: BIO FOVX -15 +15 : Defines horizontal FOV from -15 to +15 degrees. BIO FOVY -12 +12 : Defines vertical FOV from - 12 to +12 degrees.
BIO STPX STPY step_x step_y	Angular steps in horizontal (STPX) and vertical (STPY) di- rections. The total field-of-view is therefore scanned by a rectangular array with FOVX/STPX sampling points hori- zontally and FOVY/STPY sampling points vertically.
BIO LEFT RIGHT zk	Specifies the zoom/multi-configuration position repre- senting the left or right eye, respectively. Requires that the optical system is a zoom/multi-position system. Example: BIO LEFT z1: Position 1 is taken as the left eye. BIO RIGHT z2: Position 2 is taken as the right eye.
BIO FACT scale_factor	The scale factor converting chief ray differences at the dis- play into angular aberrations. Since scale_factor is constant for all viewing angles, a linear (perfect) optical system is assumed as a reference.

Biocular analysis. FOV : Plot bi

## **Example:**

An example system showing the use of the biocular option is found in the examples directory  $i\$  and  $i\$  and  $i\$  biocular biocular. t, as shown in Fig. 14.17. This is a zoom system with two positions, each position representing the left and right eye respectively. The left eye pupil is decentered at X = -32mm, the right eye pupil is decentered at X = +32mm, giving a total pupil distance of a typical human body of 64mm.

The apparent field of view (FOV) is limited for both eyes because the lens diameters are limited in size (see FHY command) and therefore truncate rays at extreme  $\pm X$  viewing directions. This condition does allow a biocular view (i.e. with both eyes simultaneously) only in the central field of view, but not over the full field. The fields, seen by the left and right eye, respectively, are indicated in the field of view (FOV) plot (see BIO FOV command, and Fig. 14.18).

The convergence and divergence plots, as shown in Fig. 14.19, indicate the amount of accommodation required by the human eye to get sharp vision at various field points.



Figure 14.17: Biocular system with left and right eye modelled in a zoom configuration. Here shown as a 3D wire grid view.

# **14.2** Diffraction Analysis

## 14.2.1 Diffraction Modulation Transfer Function (MTF)

The diffraction Modulation Transfer Function (MTF) takes into account the extended nature of objects. It is a measure of the accuracy with which different frequency components are reproduced in the image. By default the sine wave MTF is calculated. Note, that the accuracy of the MTF calculation also depends on the density of the ray grid going through the system. Check NRD. The MTF is always calculated for the current zoom position. Use POS command to select a different position.

	1
	Plot Modulation Transfer Function versus:
	FRE = spatial frequency
	FLD = fields (default)
MTF FRE FLD DEF [NUM]	DEF = defocus
	The optional parameter NUM gives a numerical table instead of
	a plot.
MTFA [fij wij zi]	
	Calculates mean value of sagittal and tangential MTF at the
	specified field points (fij), wavelengths (wij) and
	zoom position zi. Produces numerical output only. MTF is
	computed at spatial frequency defined by the MFR command
	(see below). The resulting MTF values are in the range between
	0 and 1. When used as a function in UGR or optimization, only
	one field or zoom position can be specified.
	continued on next page

continued from previous page	
MTFS [fij wij zi]	Calculate MTF in sagittal direction at specified field points (fij), wavelengths (wij) and zoom position zi. Pro- duces numerical output only. MTF is computed at spatial fre- quency defined by the MFR command (see below). The result- ing MTF values are in the range between 0 and 1. When used as a function in UGR or optimization, only one field or zoom position can be specified.
MTFT [fij wij zi]	Calculate MTF in tangential (meridional) direction at specified field points (fij), wavelengths (wij) and zoom position zi. Produces numerical output only. MTF is computed at spatial frequency defined by the MFR command (see below). The resulting MTF values are in the range between 0 and 1. When used as a function in UGR or optimization, only one field or zoom position can be specified.
MTF2D [fi zi max_freq]	Plot 2-dimensional MTF at specified field point fi and zoom position zi for a maximum spatial frequency max_freq. MTF2D without any parameter uses field1, zoom position 1.
MFR max_freq	Maximum spatial frequency used in MTF analyses vs. spatial frequency. It is given in Lp/mm for focal systems, in Lp/mrad for afocal systems. See also MFRF which defines the maximum frequency for MTF vs. field analyses.
MFRF max_freq_field	Maximum spatial frequency used in MTF analyses vs. field. It is given in Lp/mm for focal systems, in Lp/mrad for afocal systems. See also MFR which defines the maximum frequency for MTF vs. frequency analyses.
MFRD max_freq_defocus	Maximum spatial frequency used in MTF analyses vs. defocus. It is given in Lp/mm for focal systems, in Lp/mrad for afocal systems.
IFR frequency_increment	Increment in frequency (in Lp/mm for focal systems, in Lp/mrad for afocal systems). The default id MFR/20.
AF'R autofocus_frequency or MFRA autofocus_frequency	Spatial frequency used in autofocus option. It is given in Lp/mm for focal systems, in Lp/mrad for afocal systems

The calculation of the modulation transfer function follows the treatment of Malacara [33]

$$\hat{H}(f_x, f_y) = \iint_{-\infty}^{+\infty} \hat{P}(x, y) \hat{P}^* \left( x - \lambda R f_x, \ y - \lambda R f_y \right) dxdy$$
(14.30)

where R is the reference radius and  $(f_x, f_y)$  are the spatial frequencies in either x- or y-direction. Complex quantities are indicated by carets  $\hat{}$  on the corresponding symbols.  $\hat{P}(x, y)$  is the pupil function defined by



Figure 14.18: Biocular field of view example.

$$\hat{P}(x,y) = A(x,y)e^{ik \cdot W(x,y)}$$
(14.31)

where W(x, y) is the wavefront deformation, A(x, y) is the amplitude of the wave and (x, y) are the coordinates in the exit pupil. Thus, the pupil function gives the variation in amplitude and phase across the exit pupil of the system. The phase is deduced from the wavefront aberration and the amplitude is derived from the intensity of each ray<sup>2</sup> across the exit pupil of the system. We also note the relation of amplitude and intensity response

$$I(x,y) = [A(x,y)]^2$$
(14.32)

In almost all textbooks on optics, a uniformly illuminated pupil is assumed and since for this condition A(x, y) and I(x, y) are constant (unity) at every point within the aperture, it can be omitted. However, when the transmission property of the pupil is disturbed (e.g. by obstructions of the pupil or by apodization), the amplitude factor will accurately model these effects.

We can now write the integral explicitly

$$\hat{H}(f_x, f_y) = \iint_{-\infty}^{+\infty} \overline{A} \cdot e^{ik \cdot W(x,y)} e^{-ik \cdot W(x - \lambda R f_x, y - \lambda R f_y)} dx dy$$
(14.33)

with

$$\overline{A} = A(x, y) \cdot A(x - \lambda R f_x, \ y - \lambda R f_x)$$
(14.34)

$$k = 2\pi/\lambda \tag{14.35}$$

<sup>&</sup>lt;sup>2</sup>In this context we mean the apparent intensity of rays passing the system at different pupil coordinates (x, y). Intensity variation across the pupil occurs if the system exhibits varying transmission as a function of pupil coordinate (for example in systems with high numerical aperture) or if the source itself does not emit uniformly over spatial coordinates (e.g. apodization in laser applications).



Figure 14.19: Biocular convergence/divergence example.

The integral of equation 14.33, when normalized with respect to its value at  $f_x = f_y = 0$ , is called the *optical transfer function* (OTF). It represents the convolution of the pupil and the laterally sheared image of it. Thus, the frequency response  $\hat{H}(f_x, f_y)$  for incoherent illumination, apart from a constant factor, is the auto-correlation function of the pupil function. The optical transfer function is a complex quantity, its real part is called the modulation transfer function (MTF), the imaginary part is the phase transfer function (PTF).

### **Square Wave MTF :** (reserved for future releases)

The square wave response is calculated by resolving the square wave into its Fourier components and taking the sine wave response to each component:

$$S(v) = \frac{4}{\pi} \left[ M(v) - \frac{M(3v)}{3} + \frac{M(5v)}{5} - \frac{M(7v)}{7} + \dots \right]$$
(14.36)

with:

S(v) = square wave MTF

M(v) = sine wave MTF

v = spatial frequency

## **14.2.2** Point Spread Function (PSF)

The diffraction point spread function (PSF) describes the intensity of the diffraction image formed by the optical system of a single point source in the object space. The point spread function is computed from the wavefront in the exit pupil of an optical system by a double Fourier integral as given in Eq. 14.39. Aperture obstructions and non-uniform illumination of the aperture (apodization) are correspondingly taken into account. In case of polychromatic analysis, the monochromatic PSF's are integrated over the wavelengths according to the assigned wavelength weights.



Figure 14.20: Diffraction PSF in perspective view.

The amplitude distribution A(x, y) in the exit pupil and the corresponding wavefront aberration W(x, y) define the complex pupil function P(x, y). The normalized coordinates in the exit pupil are (x, y).

$$P(x,y) = \begin{cases} A(x,y)e^{2\pi j \cdot W(x,y)/\lambda} \\ 0 \end{cases}$$
(14.37)

The pupil function P is zero outside the pupil. The intensity distribution I(x, y) in the exit pupil is given by

$$I(x,y) = [A(x,y)]^2$$
(14.38)

The diffracted irradiance  $|h(u, v)|^2$  of a point-source object in the image plane with coordinates (u, v) is well approximated by

$$|h(u,v)|^{2} = \frac{\left[\iint_{-\infty}^{+\infty} P(x,y)e^{-2\pi j(x \cdot u + y \cdot v)} dx dy\right]^{2}}{\left[\iint_{-\infty}^{+\infty} P(x,y) dx dy\right]^{2}}$$
(14.39)

#### 14.2.2.1 Patch Size

A Fast Fourier Transform (FFT) is used to compute the integral in Eq. 14.39. Due to the unit transformation properties of the Fourier Transform, there is a relation between the sampling in the exit pupil of the optical system (defined by the ray grid, see NRD command) and the sampling period in the image plane. Thus, the computed area in the image plane is a function of three parameters, the sampling period in the exit pupil, the reference wavelength and the numerical aperture of the optical system. The default sampling in the exit pupil is a grid of 32 x 32 rays (NRD = 32). The maximum patch size in the image plane which can be calculated is then determined by

$$x_{image} = \frac{\lambda N_p}{2 \cdot \sin(u')} \tag{14.40}$$

with :

- $\lambda$  = wavelength in  $\mu m$
- u' = numerical aperture in image space
- $N_p$  = number of sampling points across pupil (see NRD command)

If necessary, the maximum allowed patch size can be increased by increasing NRD (number of rays across diameter). Image patches smaller than the default value (i.e. calculated by Eq. 14.40) can be freely specified.

Another technique for the computation of the PSF is the direct integration of the complex pupil function (Huygens). This method allows direct specification of the image patch, however, it is computing intensive. It is therefore only available for the cross sectional PSF in two orthogonal sections (see PSF\_XY command).

	Calculate and	plot diffraction point spread function	
	(PSF). The parameter are:		
	PSF VIE:	perspective plot of the PSF	
	PSF GRY:	gray level plot of PSF	
	PSF TRU:	pseudo true-colour plot of PSF. The	
		colour components, contributing to the	
		polychromatic PSF are coded into a	
		rgb-model to give an impression of	
		chromatic aberrations in the PSF.	
	PSF FAL:	"false" colour PSF. The intensity of the	
		PSF is coded into a rgb-model. Blue	
		colour represents low intensities, red	
PSF fk [zk]		colour represents high intensities.	
[VIE GRY CON XY ZOO	PSF CON:	contour plot of PSF	
norm log] [img_size]	PSF XY:	cross sectional plots (in X- and Y-	
		direction)	
	PSF ZOO:	zoom (resample) the PSF to a desired	
		image area.	
	norm:	can be used in conjunction with PSF	
		VIE and normalizes the PSF to unity,	
		independent of the actual value of the	
		Strehl-ratio.	
	log :	plots the PSF on a logarithmic scale.	
	img_size:	Size of the image patch. See sect.	
		14.2.2.1 for restrictions on patch size.	
PSF FF patch [FIL			
file_name] [?]	Full field PSF.	The gray-scale PSF is computed at nine	
	discrete field po	oints within the maximum field. See also	
	section 14.2.5 f	for a detailed description.	
PSF DF [img_size   fij]			
	Diagonal field l	PSF. The PSF is computed at all specified	
	field points and	displayed in a single gray-coded bitmap.	
	See also section	n 14.2.4 and Fig. 14.21.	
		continued on next page	

continued from previous page	
PSF fk [zk] [img_size] FIL file_name	Write PSF intensity data to file file_name. The file written is a ASCII-file with 4*NRD columns and rows.

## 14.2.2.2 Exporting PSF-Data

Intensity distributions resulting from point spread function (PSF) calculations may also be written to a file. The file format is plain ASCII as described in sect. 32.12.

PSF fk [zk] [img_size] FIL	Write PSF intensity data to file file_name. The
file_name	file format is either ASCII or Excel, defined by
	the file extension (*.txt or *.dat for ASCII,
	*.xls for Excel). The number of rows and
	columns is 4*NRD, i.e. NRD 32 will write a 128
	x 128 matrix. See sect. 32.12 for a description of
	the file format.

## 14.2.3 PSF Diameter in X and Y, Ellipticity

The diameter of a PSF can be calculated along two slices, in x- and y-direction. The intensity level at which the diameter is calculated can be freely defined. By default this level is at the  $1/e^2$  intensity.

PSD fi zi [threshold]	Calculates diameter of PSF for a given field fi and zoom position zi. By default, the diameter is mea- sured in the Y-direction and is determinated at a cer- tain intensity level, defined by the threshold, a value between 0 and 1. threshold is optional with a default value = $1/e^2 = 0.135$ . Example: psd f1 z3 0.135 Calculate the diameter of the PSD in Y-direction at an intensity threshold of 0.135
PSDX fi zi [threshold] or PSDY fi zi [threshold]	Calculates diameter of PSF in X-direction or in Y- direction for a given field fi and zoom position zi. The diameter is determinated at a certain intensity level, defined by the threshold, a value between 0 and 1. threshold is optional with a default value = $1/e^2 = 0.135$ .
PSE fi zi [threshold]	Calculates the ellipticity of the PSF for a given field fi and zoom position zi. The ellipticity of the PSF is defined as the ratio of x-diameter (PSDX) and y-diameter (PSDY) at the (optional) threshold- intensity, a value between 0 and 1. The PSE of a perfect (round) PSF is 1.

## 14.2.4 Diagonal Field PSF

It is sometimes desirable to simultaneously show the dependency of the PSF over the whole field of view instead for a single object point only, as (for example) provided by the PSF GRY command. To

accomplish this, the PSF is computed at all field points specified in the field configuration (page 44) and displayed in a single bitmap image. Usually, for rotationally symmetric systems, fields are selected from the axis (center of field) to the maximum field, the diagonal of the x- and y-fields. Hence the name *diagonal-field* PSF. However, this option is also well suited for analysis of non-rotationally symmetric systems if the field points are appropriately specified in x- and y-directions.

PSF DF [patch] [FIL file_name] [?]	Calculates PSF at discrete field points arranged along the diagonal of the full-field circle. The patch size (patch) is the area at the image plane. If omitted or 0, patch is calculated automati- cally on the basis of NRD, wavelength and nu- merical aperture of the system. The resulting bitmap image may be saved to a bitmap file where the file extension defines the file format. For example, *.bmp = Windows bitmap, *.pcx = ZSoft PC Paintbrush, *.png = Portable Network Graphics. Example:
	Example: psf df 0.05 fil c:\psf.bmp



Figure 14.21: Diagonal field PSF as gray-coded bitmaps, using the PSF DF command.

## 14.2.5 Grid Field PSF

This option calculates the diffraction PSF at discrete field points arranged in a grid and displays the resulting PSF's as gray-scale images in a single bitmap image. Note, however, that the PSF's are always calculated including all wavelengths and corresponding weights whereas only the display is gray-scale.

This calculation takes the maximum (full) field circle as defined in the field configuration (page 44) and fits a square grid of field points into this circle. The field can be divided into grids defined by 3x3 and 5x5 field points. Currently the grid numbers can only be defined from the option dialog (use PSF FF ? command to invoke the dialog).

PSF FF [patch] [FIL file_name] [?]	Calculates PSF at discrete field points arranged in a grid enclosed in the full-field circle. The patch size (patch) is the area at the image plane. If omitted or 0, patch is calculated automati- cally on the basis of NRD, wavelength and nu- merical aperture of the system.
or PSF GRD [patch] [FIL file_name] [?]	The resulting grid image may be saved to a bitmap file where the file extension defines the file format. For example, *.bmp = Windows bitmap, *.pcx = ZSoft PC Paintbrush, *.png = Portable Network Graphics.
	Example: psf grd 0.05 fil c:\psf.bmp

## **Example Commands:**

psf ff	Calculates PSF's on a 3x3 field grid with automatic scaling of image area (patch).
psf ff ?	Invokes a dialog box for editing parameters
psf ff 0.05	Calculates PSF's on a 3x3 field grid with fixed scaling (0.05mm) of image area (patch)
psf ff 0.05 fil 'c:\temp\psf.bmp'	Calculates PSF's on a 3x3 field grid with fixed scaling (0.05mm) of image area and writes the grid image to file c:\temp\psf.bmp. Note that the apostrophes are only required in case of blanks in file name or folder name.

Two examples of a full-field (grid) PSF are given in Fig. 14.22





Figure 14.22: Full field (grid) diffraction PSF. Left: 3x3 field grid with X/Y field coordinates, right: 5x5 field grid.

Rendering of the PSF-images at each grid point may be reversed in case of systems with intermediate images. This option is currently only available via the option dialog box (i.e use command PSF GRD ?).

## 14.2.6 X/Y Cross Sections of PSF

Plots cross sections of the PSF in both X-section (sagittal) and Y-section (tangential) for each field specified. The PSF is referred to the coordinates of the chief ray at the reference wavelength. For afocal systems (see AFO YES), units are measured in milli-radians (mrad).



Figure 14.23: X/Y cross section of PSF

## 14.2.7 Extended Objects (Fourier Method)

This section deals with image analysis of spatially coherent and spatially incoherent objects of finite extension. It is based on Fourier theory and accounts for the limited frequency response, aberrations and diffraction effects of real optical systems on image formation. The user should be familiar with Fourier Optics (see for example the excellent book by J.Goodman, Ref. [17]) before meaningful conclusions can be drawn from this analysis.

When we speak of extended objects, or alternatively and equivalently of extended images, the spatial extension of the object area must be small so that the optical transfer function (OTF) of the optical systems does not change noticeably. Thus, for a selected field point the object of interest must be confined to the region for which the OTF remains stable.

EIMD	fk	wk	obj_type	ext_x	ext_y	?	fil	bitmap_file	
									continued on next page

continued from previous page Extended object/image, based on diffraction analysis. Uses Fourier techniques to calculate the image of an extended object at field number fk and wavelength number wk. obj\_type specifies the object type from a set of predefined objects, which can be CIR = top hat, circularELL = top hat, elliptical REC = top hat, rectangular,  $(ext_x, ext_y)$  define the width in X/Y-direction) GAU = Gaussian profile, (ext\_x, ext\_y define the  $1/e^2$  diameters) GRA = grating, (ext\_x defines the grating period) PIN = double pinhole, (ext\_x, ext\_y define the pinhole X/Y-separations) ? The question mark is optional and invokes a dialog box for editing parameters. fil bitmap\_file specifies a RGB-bitmap file as object. Supported file formats are BMP, PCX, PNG and INT. The physical extensions of the bitmap (ext\_x, ext\_y) must always be smaller than the maximum allowed object extension (see also Fig. 14.24 and the discussion below. Otherwise increase NRD). Examples: eimd f3 w2 rec 0.1 0.05 Calculates imaging of a rectangular object (width = 0.1 mm, height = 0.05 mm) at field number 3 and wavelength number 2. eimd f3 w2 fil c:\mybitmap.bmp A bitmap is used as object. eimd ? Invokes a dialog box for editing all parameters.

The extended images calculated by this option may also be exported to files. Currently the INT-format (see section 32.11) and a "raw" format are available. The data in the "raw" file span the numerical range between 0 and 1. Export to INT or "raw" files, however, is only possible from the option dialog of an extended image window.

Since the algorithm used for calculating the extended image is based on Fast Fourier Transforms (FFT), the physical size of the object array respectively the maximum allowed size of the extended object  $x_{object}$  cannot be freely chosen. Due to the unit transformation of the Fourier Transform, the sampling in the exit pupil (see NRD command) and the sampling in the object/image plane are closely related. Thus, the maximum extension x of the object/image area is defined by the number of sampling points in the pupil ( $N_p = NRD$ ), the wavelength used and the numerical aperture (sin(u)).

$$x_{max.object} = \frac{\lambda N_p}{2 \cdot sin(u)}$$

$$x_{max.image} = \frac{\lambda N_p}{2 \cdot sin(u')}$$
(14.41)

Therefore, a denser aperture sampling (larger NRD) must be chosen to increase the maximum allowed object/image patch.

The object extensions must not be confused with the maximum array extensions, which are defined by Eqs. 14.41. Fig. 14.24 shows the definition of object extensions, which must always be smaller than the array dimensions, independently whether the structure is given in the object space or in the image space.



Figure 14.24: Extended object, definition of object extensions and array extensions.

#### Theory:

To analyse the imaging properties of extended objects (extended images) several assumptions are made. All imaging elements of an optical systems are combined in a single "black box" whose optical interfaces consist of the planes containing the entrance and exit pupils (see Fig. 14.25). It is furthermore assumed that the passage of light between the entrance and exit pupils is completely described by geometrical optics (i.e. using rays).

*All* diffraction effects are associated with either of these pupils and diffraction which might occur inside the optical system (the black box) is ignored. This point of view is the major difference to the physical optics beam propagation approach (see chapter 16, page 321), which does account for these effects, however, at the expense of increased computing overhead.

In describing the underlying theory of extended source imaging we shall follow the excellent description of Fourier optics by Goodman [17]. In this section only a condensed summary is given. The reader interested in a more complete treatment may wish to consult Goodman's book.



Figure 14.25: Generalized black-box model of an optical system.

The image amplitude  $U_i(u, v)$  is represented by the superposition integral

$$U_i(u,v) = \iint_{-\infty}^{\infty} h(u,v) U_0(\xi,\eta) d\xi d\eta$$
(14.42)

where h(u, v) is the (complex) amplitude in the image plane in response to a point-source object at coordinates  $(\xi, \eta)$  and  $U_0(\xi, \eta)$  is the amplitude distribution of the object. For an ideal (diffraction limited) system, h is simply the Fraunhofer diffraction pattern of the exit pupil, centered at coordinates  $u = m \cdot \xi$ ,  $v = m \cdot \eta$  where m is the magnification. See also section 14.2.2, in particular Eq. 14.39, for computation of h.

In the general case, for an aberrated system, we can regard the image as being a convolution of the image predicted by geometrical optics with an impulse response that is the Fraunhofer diffraction pattern of an aperture with amplitude transmittance P, where P is defined as

$$P(x,y) = A(x,y)e^{jkW(x,y)}$$
(14.43)

W(x, y) is the wavefront aberration as predicted by the optical path difference (OPD) with respect to a reference sphere and A(x, y) is the relative amplitude in the exit pupil. Eq. 14.43 is equivalent to the optical transfer function (OTF) for the coherent case.

Using Fourier optics, we define the frequency spectra of the components

$$G_0(f_x, f_y) = \iint_{-\infty}^{\infty} U_0(u, v) e^{-2\pi j (f_x u + f_y v)} du dv$$
(14.44)

$$G_i(f_x, f_y) = \iint_{-\infty}^{\infty} U_i(u, v) e^{-2\pi j (f_x u + f_y v)} du dv$$
(14.45)

$$H(f_x, f_y) = \iint_{-\infty}^{\infty} h(u, v) e^{-2\pi j (f_x u + f_y v)} du dv$$
(14.46)

Applying the convolution theorem, it follows directly that

$$G_i(f_x, f_y) = H(f_x, f_y)G_0(f_x, f_y)$$
(14.47)

where we have expressed the effects of imaging in the frequency domain.

#### The coherent case:

For coherent imaging, the optical transfer function  $H(f_x, f_y)$  can be directly related with the amplitude transmittance P

$$H(f_x, f_y) = P(\lambda z_i f_x, \lambda z_i f_y)$$
(14.48)

where  $z_i$  is the distance from the exit pupil to the image plane.

#### The incoherent case:

$$H(f_x, f_y) = \frac{\mathcal{F}|h(u, v)|^2}{\iint |h(u, v)|^2 du dv}$$
(14.49)

which is equivalent to Eq. 14.46, except that the phase information of the complex amplitude of the point-source image is rejected. H now specifies the complex weighting factor applied by the system to the frequency component at  $(f_x, f_y)$ . Note that the modulus |H| is known as the modulation transfer function (MTF). See also section 14.2.1, where the autocorrelation method is used to calculate |H|.

#### **Operator Notation:**

Both coherent and incoherent imaging can also be expressed in operator notation, where  $\mathcal{F}$  denotes Fourier Transform and  $\mathcal{F}^{-1}$  denotes the inverse Fourier Transform.

Coherent case:

$$U_{i}(u,v) = \mathcal{F}^{-1} \left[ \mathcal{F} \left[ U_{0}(\xi,\eta) \right] P(x,y) \right]$$
(14.50)

Incoherent case, without explicit notation of the normalization integral in Eq. 14.49:

$$U_i(u,v) = \mathcal{F}^{-1} \left[ \mathcal{F} \left[ U_0(\xi,\eta) \right] \mathcal{F}^{-1} \left[ |h(u,v)|^2 \right] \right]$$
(14.51)

### 14.2.8 Knife Edge Function (KEF)

The knife edge function, also called "edge spread function" or "slant edge function", calculates the response of a "sharp edge" in the image plane.

KEFS fk	Compute the width of the knife edge function (KEF) in the sagittal di- rection at field fk. Typically, the width is defined by the 10% and 90% intensity points of the KEF. See the KEFL and KEFH commands to set the intensity levels of the KEF.
KEFT fk	Compute the width of the knife edge function (KEF) in the tangential direction at field fk.
KEFL I_low I_high	Set the low and high intensity levels for calculating the width of the knife edge function. The levels must be entered in percent (%). Default values are $I_{low} = 10$ , $I_{high} = 90$ .
KEFH I_high	Set the high intensity level for calculating the width of the knife edge function. The level must be entered in percent (%). Default value is $I_high = 90$ .
	continued on next page

continued from previous page	
PLO KEF fk [?]	Plot knife edge function (KEF) in sagittal and tangential directions at
	field fk. The optional question mark invokes a dialog box for editing
	plotting and calculation parameters. Specify a field number fk, other-
	wise the field from a previous calculation will be used (default $fk = 1$ ).

## 14.2.9 Encircled / Ensquared Energy (Diffraction based)

The encircled energy is the fraction of total energy in the point image enclosed within a circle or square of a given size. This type of analysis is particularly useful on a detector array with square pixels to determine which fraction of total energy is contained within the size of one pixel.

Encircled/ensquared energy calculations are based on integration of the diffraction point spread function (PSF) referred to the centroid of the diffraction PSF.

The accuracy of the calculation depends on the ray grid (see NRD, number of rays across diameter). The larger NRD (i.e. the denser the rays in the pupil are) the more accurate results can be obtained.

ECE fk diam	Compute encircled energy within a diameter (diam) at field fk. Calculation is referred to the center of gravity of the PSF function. See also the EQE command below.
EQE fk diam	Compute ensquared energy within a diameter (diam) at field fk. Calculation is referred to the center of gravity of the PSE function
	fation is referred to the center of gravity of the FSF function.
PLO ECE EQE fk	Plot encircled or ensquared energy within diameter (diam) at field fk.
diam [NUM] [?]	Calculation is referred to the center of gravity of the PSF function. The
	optional question mark invokes a dialog box for editing plotting and cal-
	culation parameters. Specify a field number fk, otherwise the field from
	a previous PSF or ECE calculation will be used (default $fk = 1$ ). The
	parameter NUM outputs encircled/ensquared energy data numerically in
	the text window. Two curves will be plotted for <i>encircled</i> energy and <i>en-</i>
	<i>squared</i> energy separately. The ensquared energy curve is always higher
	than the encircled energy curve.

### Notes:

The encircled/ensquared energy is computed from the diffraction point spread function (PSF). First, the center of gravity of the PSF function is searched and from that point integration over the diameter is started. In case of non-symmetric PSF-distributions, however, the center of gravity will not be in the center of the computational FFT-grid and the integration range may be smaller than computed in the FFT-grid. The corresponding encircled energy plot will then report a smaller integration range than requested.

## 14.2.10 Strehl Ratio

The Strehl ratio (also called Strehl definition) is the ratio of the peak value of the PSF to the peak of the PSF for an equivalent ideal (*unaberrated*) system. The Strehl ratio is a number between 0 and 1, where a Strehl ratio 1 corresponds to the ideal system.

STREHL [zij fij	Numerical output of Strehl ratio for zoom positions
wij]	zij fields fij and wavelengths wij
PLO STREHL FLD	Plot Strehl ratio vs. field
PLO STREHL LAM [y-min	Plot Strehl ratio vs. wavelength. The Y-plot range can
y-max]	be adjusted by the optional parameters y-min, y-max
	(range 0 - 1).

The Strehl ratio is computed from the complex pupil function P(x, y) by

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$$STREHL = \frac{\left[\iint P(x,y) \, dx \, dy\right]^2}{\left[\iint A(x,y) \, dx \, dy\right]^2} \tag{14.52}$$

where the integration takes place over the exit pupil with coordinates (x, y). A(x, y) is the amplitude distribution in the exit pupil as defined in Eq. 14.37.

It is interesting to note that for systems with small aberrations the Strehl ratio is directly related to the variance of the wavefront  $(\triangle W)^2$ 

$$STREHL \sim 1 - \left(\frac{2\pi}{\lambda}\right)^2 (\Delta W)^2$$
 (14.53)

## 14.2.11 Wavefront Aberration (Optical Path Difference)

The wavefront aberration (or optical path difference) is the departure of the actual wavefront from the reference sphere. The reference sphere has its center of curvature at the geometrically perfect point image. There is some freedom in choosing the radius of the reference sphere. By default, OpTaliX locates the reference sphere in the exit pupil of the optical system. For the purpose of calculating the wavefront, the center of the reference sphere is always at the location of the chief ray in the image plane. Note, that in other diffraction calculations (e.g. MTF) the minimum variance of the wavefront for all wavelengths is chosen.

Wavefront calculations always include phase changes introduced by coatings on optical surfaces, if applied. This effect is normally small, however, may noticeable affect wavefront on systems with steep incidence angles (e.g. wide-field systems or high numerical aperture systems). See also section 20.6.

WAV [TLT] [ fij   wij   zij ]	Evaluate RMS wavefront aberration at fields fij, wavelengths wij or zoom positions zij. Output is given numerically. By default wavefront tilt is not sub- tracted. The TLT option, however, allows subtraction of wavefront tilt.
WAVZ [ fij   wij   zij ]	Evaluates RMS wavefront aberration as in the WAV command given above, however, allows subtraction of Zernike wavefront components like defocus, astigmatism, etc. Any order of Zernike terms is permitted. Use the ZWACT command (page 150 to define the Zernike terms to be subtracted prior to evaluating RMS wavefront aberration. Numerical output only.
PLO WAV [ FLD   LAM ]	Plot wavefront aberration vs. field (FLD) or wavelength
[TLT] [zk]	(LAM). The default is FLD. A plot scale (in microns) is queried in a dialog box. Choosing plot scale 0 will au- tomatically adjust the scale to the maximum wavefront aberration at each field/wavelength/zoom position. By default wavefront tilt is not subtracted. The TLT option, however, allows subtraction of wavefront tilt.
OPD [ fij   wij   zij ] rel_apeX rel_apeY	Optical path difference (in mm) along a single ray, re- ferred to the chief ray.
OPDW [ fij   wij   zij ] rel_apeX rel_apeY	Optical path difference along a single ray, expressed in wave units at the reference wavelength.



Figure 14.26: Wavefront aberration, shown for one discrete field point.

## 14.2.12 Conrady D-d Chromatic Aberration

ration is given in section 14.2.12, page 287).
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In achromats or apochromats, correcting the axial chromatic aberration for paraxial rays (for example see SSR command) does not mean that the longitudinal (axial) aberration vs. wavelength is also
corrected for marginal rays. The variation of spherical aberration with wavelength is called chromatic spherical aberration, or spherochromatism.

The Conrady method [9] of controlling spherochromatism is defined as

$$DMD = \sum_{i=0}^{k} (D-d) \cdot (n_F - n_C)$$
(14.54)

where D is the optical path of a ray through the aperture center and d is the optical path for a marginal ray. Often the best choice is to correct the chromatic aberration at an aperture height  $y_ape = 0.7$ .

#### 14.2.13 Single-Path Interferogram

Simulates an interferogram as it is expected from the wavefront deformation in a typical interferometer setup. Note that this analysis does not simulate a "true" two-path interferometric setup where two wavefronts physically interfere. It merely relates the optical path difference (wavefront) to the reference wavelength and displays the amount of constructive/destructive interference. Simulation of interferometric setups with two paths (arms) is discussed in the next section (dual-path interferogram).

The analysis accounts for vignetting and special apertures (central obstructions, spider, etc.). A tilt of the (interferometer) reference plane may be introduced to control the orientation of the fringes.



Figure 14.27: Interferogram, computed from wavefront aberration at one discrete field point.

#### **Command syntax:**

IFG field_number	Compute the interferogram from the wavefront deformation at	
	the reference wavelength.	

#### 14.2.14 Dual-Path Interferogram

This option calculates the wavefront of two separate configurations and superimposes it according to the law of constructive/destructive interference. The output signal is therefore similar to that seen in a typical interferometer.

INT2P sk [?]		
	Two-path interferogram. Traces two paths in an interferometric	
	setup and superimposes the resulting wavefronts. Based on construc-	
	tive/destructive interference of the two wavefronts, the interferometer	
	output is simulated and displayed. The two paths must be defined in a	
	zoom/multi-configuration setup containing at least two positions. sk	
is the target surface at which the superposition of the two wavefront		
	analyzed. The optional question mark opens a dialog box for editing	
	more parameters.	

Simulation of two separate paths in an interferometer requires a zoom/multi-configuration setup with at least two positions. An example (Mach-Zehnder interferometer) is shown in Fig. 14.28. See also the examples library in the interferometer section.

The aperture of the target surface defines the area over which the interferogram is constructed. The aperture extension (e.g. CIR, or REY, or ELY) of the target surface should be at least the size of the expected beams to cover the full interferogram.



Figure 14.28: Example of a Mach-Zehnder interferometer with a test piece in arm B. Non-sequential surfaces and zoom configurations create the interferometer. The surface error of the test piece is described by a Zernike deformation.

## 14.3 Gaussian Beams

*Gaussian beams*, such as the laser beam, are highly directional and have a spatially non-uniform (radially symmetric) intensity distribution. Its Fourier transform is also a Gaussian and it remains Gaussian at every point along its path of propagation through the optical system. The Gaussian has no obvious boundaries, so the commonly agreed definition of the size of Gaussian is the radius at which the intensity has decreased to  $1/e^2$  of its value on the axis.

	BEA [wi	j   zij  ?]
		Gaussian beam analysis at wavelength numbers ij, zoom positions ij. The reference wavelength is used if no wavelength range (wii) is given
		The input beam has a gaussian intensity profile and starts at the object surface i.e. the
		waist of the beam is assumed at the object surface. Analysis requires proper setting
		of waist size (see MDV - MDV below)
		The optional question mark invokes a dialog box for editing of MPX MPX 7MX
		The optional question mark invokes a dialog box for cutting of WRA, WR1, ZWA,
		ZWI, RCA, RCI allu MZ.
	WRX X_rad	
		Waist radius (in mm) in X-direction at object surface, respectively relative to surface
		sk at zoom position zij zk and wavelength(s) wij wk. Only one parame-
		ter may be given in a command, either $x_rad$ or $sk   zk   wk$ . The optional surface
		parameters sij sk, zij zk and wij wk (without x_rad) are only ap-
		plicable when WRX is used as a function. Examples:
		wrx 0,005 ! waist X-radius at object plane is 0.005mm
		wry s6 1 returns waist X-radius at surface 6 in buffer for use in LIDG or optimiza-
		tion
		$\frac{1}{2}$
		matter 2 and wavelength 2 in buffer for use in LIDC or entimization. Note that the
		position 5 and wavelength 2 in burlet for use in ODG of optimization. Note, that the
		2 k parameter is obligatory for zoomed systems.
	WRY y_rad	[sk  wij zij]
		Waist radius (in mm) in Y-direction at object surface, respectively relative to surface
		sk at zoom position zk and wavelength(s) wij   wk. Only one parameter may be
		given in a command, either $y_rad$ or $sk   zk   wk$ . The optional surface parameters
		sij sk, zij zk and wij wk (without y_rad) are only applicable when
		WRY is used as a function.
		Examples:
		wry 0.005 ! waist Y-radius at object plane is 0.005mm
		wry s6 ! returns waist Y-radius at surface 6 in buffer for use in UDG or optimiza-
		tion.
		wry s6 z3 ! same as above, but returns waist Y-radius at surface 6 for zoom
		position 3 in buffer for use in UDG or optimization. Note, that the zk parameter is
		obligatory for zoomed systems.
Ì	RCX wave_r	rad_x [sk  wii zii]
		Radius of curvature of wavefront in x-direction at object plane, respectively rel-
		ative to surface sk at zoom position $z_1$ $i \perp z_k$ and wavelength(s) wi $i \perp w_k$
		Only one parameter may be given in a command either wave rad or skizkiwk
		The optional surface parameters $s_1$ is $s_2$ is $s_1$ and $w_1$ is $w_2$ (without
		The optional surface parameters $5 \pm \dots \pm 5^{-}$ , $2 \pm \dots \pm 5^{-}$ , $2 \pm \dots \pm 5^{-}$ and $w \pm \dots \pm 5^{-}$ (without when we have $m = 1$ and $m = 1$ and $m = 1$ .
		wave_rau) are only applicable when NCA is used as a function.
Ц	1	

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Examples:		
rcx 0 ! wavefront X-radius of curvature at object plane is infinity.		
	rcx s6 ! returns wavefront X-radius of curvature at surface 6 in buffer for use in	
	UDG or optimization.	
	rcx s6 z3 ! same as above, but returns wavefront X-radius of curvature at sur-	
	face 6 for zoom position 3 in buffer for use in UDG or optimization. Note, that the	
	zk parameter is obligatory for zoomed systems.	
RCY wave_r	rad_v [sk  wii zii]	
	Radius of curvature of wavefront in v-direction at object plane, respectively rel-	
	ative to surface sk at zoom position $z_{1}$ , $z_{1}$ and wavelength(s) with $z_{1}$ wk	
	Only one parameter may be given in a command either wave rad or $sk   zk   wk$	
	The optional surface parameters $s_1$ $i \mid s_k \mid z_1 \mid i \mid z_k \mid and \mid i \mid i \mid w_k$ (without	
	wave rad) are only applicable when $\mathbb{RCV}$ is used as a function	
	Examples	
	rcy 1000 ! wavefront Y-radius of curvature at object plane is 1000mm	
	rcy s6   returns wavefront Y-radius of curvature at surface 6 in huffer for use in	
	UDG or optimization.	
	$r_{CV}$ s6 z3 $l$ same as above but returns wavefront Y-radius of curvature at surface	
	6 for zoom position 3 in buffer for use in UDG or ontimization. Note that the $zk$	
	narameter is obligatory for zoomed systems	
7WX z-wais	zt – v [ek  wi j zi j]	
	U contion of beam waist relative to object plane for y direction respectively relative	
	Location of beam waist relative to object plane for x-direction, respectively relative to surface $ak$ at zoom position $z_i = \frac{1}{2}  z_i ^k$ and we valength(a) $w_i = \frac{1}{2}  w_i ^k$ . Only	
	to surface SK at zoolin position $21$ $ ZK$ and wavelengin(s) $w1$ $ wK$ . Only	
	The entire all surface percentations of $\frac{1}{2}$ of $\frac{1}{2}$ and $\frac{1}{2}$ of $\frac{1}{2}$ without	
	The optional surface parameters $S_{1}$ , $J_{1}S_{k}$ , $Z_{1}$ , $J_{2}K$ and $w_{1}$ , $J_{1}W_{k}$ (without $z_{1}$ , $w_{2}$ , $w_{3}$ , $z_{2}$ , $w_{3}$ , $w_{1}$ , $w_{2}$ , $w_{1}$ , $w_{2}$ , $w_{3}$ , $w_{1}$ , $w_{2}$ , $w_{1}$ , $w_{2}$ , $w_{3}$ , $w_{1}$ , $w_{2}$ , $w_{3}$ , $w_{1}$ , $w_{2}$ , $w_{3}$ , $w_{1}$ , $w_{2}$ , $w_{2}$ , $w_{3}$ , $w_{1}$ , $w_{2}$ , $w_{2}$ , $w_{1}$ , $w_{2}$ , $w_{2}$ , $w$	
	Examples:	
	$z_{\rm WX} = 1 - 3$   X-waist is 1.3mm from object plane	
	Zwx s6 I returns X-waist position relative to surface 6 into buffer for use in IIDG	
	or optimization	
	$_{\rm ZWX}$ s 6 $_{\rm Z}$ 3 $_{\rm ZWX}$ same as above, but returns X-waist position relative to surface 6 for	
	zoom position 3 in huffer for use in LIDG or optimization. Note that the zk parameter	
	is obligatory for zoomed systems	
7WV R-MOS	- is confactly for zoomed systems.	
LWI Z-WALS	Location of beam weist relative to object plane for V direction respectively relative	
	to surface of at zoom position $z_{i}^{-1}$ $z_{i}^{-1}$ and we value $z_{i}^{-1}$ $z_{i}^{-1}$ $z_{i}^{-1}$	
	to surface SK at zoom position $21 j   ZK$ and wavelength(s) $w1 j   wK$ . Only	
	one parameter may be given in a command, entrer $z$ -waist- $y$ or $sk   zk   wk$ .	
	The optional surface parameters S1] SK, Z1] ZK and W1] WK (Without	
	z=waist=y) are only applicable when ZWY is used as a function.	
	Examples.	
	$2 \text{ wy } 1.5 \pm 1$ -waist is 1.511111 110111 00 jett plate	
	2 wy 50 ! returns 1-waist position relative to surface o into duffer for use in UDG	
	or optimization. $V_{\text{max}} = C_{\text{max}} + C_{\text{max}} +$	
	zwy so z3 ! same as above, but returns Y-waist position relative to surface 6 for	
	zoom position 5 in buffer for use in UDG or optimization. Note, that the zk parameter	
	is obligatory for zoomed systems.	
	continued on next page	

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M2	$M^2$ factor, describing the departure of real beams from the Gaussian ideal. See also Eq. 14.60. $M^2$ is the amount by which the beam waist product exceeds the diffraction limit of an ideal Gaussian beam of the same wavelength. $M^2 = 1$ for the ideal beam.		
SRX sk wi	j zij		
	Returns the Gaussian spot size in the X/Z plane at surface sk. It takes the Gaussian source parameters (such as WRX, WRY, RCX, RCY, etc.), hence they must be properly set before this function may be used. This is a function, not a command, to be used in UGR or optimization.		
SRY sk wi	j zij		
	Returns the Gaussian spot size in the Y/Z plane at surface $sk$ . It takes the Gaussian		
	source parameters (such as WRX, WRY, RCX, RCY, etc.), hence they must be		
	properly set before this function may be used. This is a function, not a command,		
CDV als set			
GDX SK WI	<b>Paturns the divergence of a Gaussian beam in the <math>X/Z</math> plane at surface <math>zk</math>. It takes</b>		
	the Gaussian source parameters (such as $MPX = MPX = PCX = CX$ at c) hence		
	they must be properly set before this function may be used. This is a function not		
	a command to be used in LIGB or optimization		
GDY sk wi	GDY sk wi ilzi i		
	Returns the divergence of a Gaussian beam in the Y/Z plane at surface sk. It takes		
	the Gaussian source parameters (such as WRX, WRY, RCX, RCY, etc.), hence		
	they must be properly set before this function may be used. This is a function, not		
	a command, to be used in UGR or optimization.		
RRX sk wi	j zij		
	Returns the Rayleigh range of a Gaussian beam in X-direction at surface sk. It		
	takes the Gaussian source parameters (such as WRX, WRY, RCX, RCY, etc.),		
	hence they must be properly set before this command may be used. This is a		
	function, not a command and may only be used in UGR or optimization.		
RRY sk wi	j zij		
	Returns the Rayleigh range of a Gaussian beam in Y-direction at surface sk. It		
	takes the Gaussian source parameters (such as WRX, WRY, RCX, RCY, etc.),		
	hence they must be properly set before this command may be used. This is a		
	function, not a command and may only be used in UGR or optimization.		

#### Mathematics:

Because of the self-Fourier Transform characteristics, complex integrals to describe the propagation of Gaussian beams are not required, since only the radius of the Gaussian ("spot size") and the radius of curvature of the wavefront change.

The variation of spot size w and wavefront radius of curvature R with distance z can be described explicitly as

$$w^{2}(z) = w_{0}^{2} \left[ 1 + \left( \frac{\lambda z}{\pi w_{0}^{2}} \right)^{2} \right]$$
(14.55)

The spot size has its minimum value at z = 0, which is equal to the beam waist  $w_0$ . The wavefront radius of curvature becomes infinity at the beam waist as illustrated in Fig. 14.29. The far-field divergence angle  $\theta$  is given by



Figure 14.29: Propagation of a Gaussian beam.

The entire beam behaviour is completely specified by any two of the four parameters  $w, w_0, R$  and  $\lambda$ . The Rayleigh range is the distance from the waist to the axial point of minimum wavefront radius of curvature

$$z_r = \frac{\pi w_0^2}{\lambda} \tag{14.58}$$

*R* has its minimum value at  $z = z_r$ . In the free space between lenses, Eqs. 14.55 and 14.56 completely describe the beam. When the beam passes through an optical interface (lens, mirror), the wavefront curvature is changed, resulting in new values for size and position of the beam waist. At the optical interface, the beam diameter does not change.

A so-called  $M^2$  factor has been introduced by Siegman[50] to describe the departure of a real beam from a Gaussian ideal beam. From Eq. 14.57 we see that the product of beam waist and far-field divergence angle is constant for a given wavelength

$$w_0\theta = \frac{\lambda}{\pi} \tag{14.59}$$

For a real beam the corresponding product can be written as

$$M^2 w_0 \theta = M^2 \frac{\lambda}{\pi} \tag{14.60}$$

Thus, the propagation of the spot size of real beams described by an  $M^2$  factor is described by the same equation as for an ideal Gaussian.

(14.57)

It has been shown by Kogelnik and Li [27] and Herloski, Marshall and Antos [20], that the propagation and transformation of anastigmatic *Gaussian beams* can be modelled by an orthogonal characteristic ABCD matrix in the paraxial domain and, furthermore, can be represented by two paraxial rays. Following the model of Arnaud [2], we choose a waist ray (tangent to the input beam at the waist) and a divergence ray (tangent to the input beam at infinity), as shown in Fig. 14.30. Recalling the equations of Kogelnik and Li, we obtain

$$w' = \sqrt{y_d^2 + y_w^2}$$
(14.61)

$$z' = \frac{y_d v_d + y_w v_w}{v_d^2 + v_w^2} \tag{14.62}$$

$$w_0 = \frac{y_w v_d - v_w y_d}{\sqrt{v_d^2 + v_w^2}} \tag{14.63}$$



Figure 14.30: Equivalent paraxial rays for modelling of Gaussian beam propagation.

#### 14.4 Fiber Coupling Efficiency

Calculation of coupling efficiency (CEF) includes apodization, clipping of the input beam, reflection losses by coated or uncoated surfaces and bulk absorption.

CEF [ ?   fi   wi ]	Calculate linear coupling efficiency (CEF). The question mark (optional) invokes a dialog box for editing proper- ties of source fiber and receiving fiber.
CEFDB [ ?   fi   wi ]	Calculate coupling efficiency in decibel instead of re- turning the linear value. See also the CEF command above.
	continued on next page

continued from previous page	
	Mode profile. Select
	GAU for Gaussian mode profile,
MPR GAU   STE   FIL	STE for step-index,
	FIL for user defined profile loaded from file (in
	preparation).
	Fiber location in either a fixed (FIX) or compen-
	sated (CMP) position.
	FIX : The fiber is in a fixed position in the lo-
	cal coordinate system of the image surface
	(see also the second form of the FLO com-
FIO FIXICMP	mand below). The location of the fiber is
	independent of the beam location
	CMP · The fiber position follows the chief ray
	This is the default mode. The fiber is on-
	timely shifted/tilted to give an entimized
	accurling officiancy
	Coupling efficiency.
гго x-bos À-bos	specify the coordinates of the (receiving) fiber position
	with respect to the local coordinate system of the image
	surface.
FSR rad_x rad_y	Fiber source radius in X- and Y-direction (in mm). El-
	liptical source profiles are specified by different values
	for the x- and y-extension. If only one value is given, the
	mode profile is assumed circular.
FSD div_x div_y	Far-field fiber source divergence. Elliptical far-fields are
	specified by different values for the x- and y-extension.
	If only one value is given, the far-field is assumed circu-
	lar.
FSA alpha_tilt	Fiber source $\alpha$ -tilt in degree. Specify the rotation angle
-	of the source fiber in the YZ plane. The rotation angle is
	defined in the local coordinate system.
FSB betatilt	Fiber source $\beta$ -tilt in degree. Specify the rotation angle
	of the source fiber in the XZ plane. The rotation angle is
	defined in the local coordinate system
FRR mode radius	Receiving fiber mode-field radius (in mm)
FRD div	Receiving noor mode nord radius (in min).
	Far-field divergence of receiving fiber (in rad).
FRA alpha_tilt	
	Receiving fiber $\alpha$ -tilt in degree. Specify the rotation an-
	gle of the receiving fiber in the YZ plane. The rotation
	angle is defined in the local coordinate system. See also
	Fig. 14.31 for a definition of signs.
FRB beta_tilt	
	Receiving fiber $\beta$ -tilt in degree. Specify the rotation an-
	gle of the receiving fiber in the XZ plane. The rotation
	angle is defined in the local coordinate system. See also
	Fig. 14.31 for a definition of signs.
FRX x-offset	
	Receiving fiber x-offset (in mm) with respect to the chief
	ray.
	continued on next page

continued from previous page	
FRY y-offset	Receiving fiber y-offset (in mm) with respect to the chief ray.
WDX wedge_angle_x	Wedge angle (cleavage angle) of the front face of the fiber in the X-direction, i.e. in the local XZ plane. The angle is measured in degree. See also Fig. 14.31 for a definition of signs.
WDY wedge_angle_y	Wedge angle (cleavage angle) of the front face of the fiber in the Y-direction, i.e. in the local YZ plane. The angle is measured in degree. See also Fig. 14.31 for a definition of signs.
FSN1 source_core_index	Source fiber, index of refraction $n_1$ of core material
FSN2 source_cladding_index	Source fiber, index of refraction $n_2$ of cladding material
FSCR source_core_rad	Source fiber, core radius in mm.
FRN1 receiver_core_index	Receiving fiber, index of refraction $n_1$ of core material
FRN2 receiver_clad_index	Receiving fiber, index of refraction $n_2$ of cladding material
FRCR receiver_core_rad	Receiving fiber, core radius in mm.
FIBS prod-spec	Specify source fiber by product (e.g. by manufacturers type number). A single command inserts all relevant op- tical data from a fiber catalogue. This option is currently only available from the menu.
FIBR prod-spec	Specify receiving fiber by product (e.g. by manufactur- ers type number). A single command inserts all relevant optical data from a fiber catalogue. This option is cur- rently only available from the menu.
TGR fft_grid	Transformation grid. Because the coupling option uses a Fast Fourier Transform (FFT), a $2^n$ transform grid must be specified. The default value of TGR = 128, but it may be adjusted to 64, 128, 256, 512 or 1024. Smaller values of TGR are not recommended, as the accuracy of the computation will be reduced (sampling density is to coarse). Note, that a change of TGR also affects NRD (number of rays across pupil diameter). The relation is TGR = 4 * NRD.
FSMM max_modes_source	Fiber source maximum modes. Limits the number of modes calculated in the source fiber. max_modes_source must be less than less than the highest number of possible modes N in that fiber (see Eq. 14.76). Enter FSMM -1 to always search for all modes possible (N).

continued from previous page	
FRMM max_modes_receiver	Fiber receiver maximum modes. Limits the number of modes calculated in the receiver fiber. $max_modes_receiver$ must be less than the highest number of possible modes N in that fiber (see Eq. 14.76). Enter FRMM -1 to always search for all modes possible (N).
MMF	Display field of a multi-mode fiber at selected modes. Opens a dialog box for editing fiber parameters. See a detailed description in sect. 14.4.3.

Notes:

- Coupling efficiency is normally computed for systems with finite object and image distances (fiber-fiber or diode-fiber applications). For systems, where the object is at infinity, the pupil will be assumed uniformly illuminated. All computations are then referred to the total energy incident upon the entrance pupil. Only for this special case, the Gaussian beam profile (e.g. from a collimated laser) must be properly set by the apodization factors PUI, PUX and PUY respectively. For finite object and image distances, apodization should be switched off (PUI=PUX=PUY=1), as the Fourier Transformation property based on the fiber mode profile already yields the correct far-field amplitude profile in the entrance pupil.
- The only approximation made in the computation method as described below is that diffraction effects that occur between entrance and exit pupil are neglected. In many cases this approximation is sufficiently accurate, but in special cases, for example when the beam is very small or when the free space in the optics is large, a diffraction beam propagation method (BPR) must be applied. The Fresnel number is a good indicator, whether CEF or BPR is appropriate. The Fresnel number N is a property of the beam semi diameter w, wavelength

 $\lambda$  and propagation distance L. It is given by  $N = \frac{w^2}{\lambda L}$ . For small Fresnel numbers (N < 1), beam propagation should be used, otherwise CEF can be used with sufficient accuracy.

The calculation of coupling efficiency (also known as insertion loss) involves components and optical systems, which collect light from a source (a laser, a fiber, etc.) and couple it into a receiving fiber. The basic problem is to account for the effects of aberrations, fiber misalignments and fiber-mode mismatch.

The coupling efficiency T is defined as the normalized overlap integral of the image field distribution U(x', y') and the mode pattern of the receiving fiber  $\psi(x', y')$ 

$$T = \left| \frac{\int \int U(x', y') \cdot \psi^*(x', y') dx' dy'}{\sqrt{\int \int U(x', y') \cdot U^*(x', y') dx' dy' \int \int \psi(x', y') \cdot \psi^*(x', y') dx' dy'}} \right|^2$$
(14.64)

where \* denotes the complex conjugate. For computational purposes, the method described by Wagner and Tomlinson [57] is applied in OpTaliX for which the overlap integral is transformed to the exit pupil of the coupling optics. The power-coupling efficiency T is then expressed as a single integral with an integrand that is the product of the complex far-field distributions of the source-fiber mode profile  $\Psi_S(\zeta, \eta)$ , the far-field distribution of the receiving-fiber mode profile  $\Psi_R(\zeta, \eta)$  and the coherent transfer function of the optical system  $L(\zeta, \eta)$ 



Figure 14.31: Definition of fiber tilts (FRA, FRB) and cleavage angles (WDX, WDY), here shown in the Y/Z plane only. The sign of the angles is in accordance to surface tilts. It follows mathematical convention, i.e. it is positive for counter-clockwise rotation and negative for clockwise rotation.

$$T = \left| \int \Psi_S(\zeta, \eta) \cdot L(\zeta, \eta) \cdot \Psi_R(\zeta, \eta) da \right|^2$$
(14.65)

where  $(\zeta, \eta)$  are the normalized coordinates in the exit pupil.  $\Psi_S$  and  $\Psi_R$  are the scaled Fourier transforms of the source and receiving fiber mode profiles  $\psi_s$  and  $\psi_r$  respectively. The coherent transfer function is expressed as  $L = exp[-ikW(\zeta, \eta)]$  where W is the wavefront aberration and  $k = 2\pi/\lambda$ . Thus, all aberrations (optical system wavefront error, fiber misalignments and mode profile mismatch) are described in the exit pupil of the optical system, allowing coupling effects to be handled in a manner consistent with accepted conventions in classical optics.

Using the quantities and relations given above, the far-field diffraction angle  $\theta$ , which is usually defined at the  $1/e^2$  intensity, must not be confused with the numerical aperture (NA) of the fiber and of the coupling optics. For multi-mode fibers the maximum angle of the beam radiated from (or accepted by) a fiber is determined by the refractive index difference between core and cladding and is defined by

$$NA = \sqrt{n_1^2 - n_2^2} = n_1 \sqrt{2\Delta}$$
(14.66)

where

$$\Delta = \frac{n_1^2 - n_2^2}{2n_1^2} \approx \frac{n_1 - n_2}{n_1} \tag{14.67}$$

and  $n_1$  is the index of refraction of the core,  $n_2$  is the index of refraction of the cladding. NA is conventionally used as a measure of that index difference.

For a single-mode fiber, not only the core-cladding index difference but also the core size (precisely the mode-field diameter) and the wavelength of the light define the angular beam spread. With this definition, about 25% of the emitted power propagates at angles larger than  $\theta$  (see also Fig. 14.32). In order to avoid substantial truncation of the beam, the lens NA must be extended beyond the emitted  $1/e^2$  far-field divergence angle  $\theta$ . The divergence angle, at which the far-field intensity has fallen to the 1% point is about 1.5 times larger than the  $1/e^2$  angle and the lens NA must be oversized by this factor for efficient coupling.



Figure 14.32: Transformation of the source profile (fiber or laser) to the entrance pupil of the optical system (not to scale). In the example shown, the numerical aperture (NA) of the coupling system matches the far-field divergence  $\theta$  of the source (which is defined at the  $1/e^2$  point). Hence, only a fraction of the emitted energy is transferred by the coupling optics, because the foot of the Gaussian field is truncated by the aperture stop of the optical system.

Assuming identical source and fiber modes (i.e. the Gaussian beams perfectly match), the theoretical coupling efficiency can be expressed as a function of the numerical aperture of the optics (NA) and the far-field divergence  $\theta$  of the fiber

$$T = \left(1 - \exp\left[-2\left(\frac{NA}{\theta}\right)^2\right]\right)^2 \tag{14.68}$$

For the above mentioned case, where  $NA/\theta = 1.5$ , the coupling efficiency is 0.978 (-0.097 dB).

#### 14.4.1 Single-Mode Fibers

Single-mode fiber applications are different to classical optical imaging in that the source fiber, coupling optics and receiving fiber comprise a coherent system. In single-mode fibers, only one mode propagates because the core size (typically  $5 - 10 \mu m$ ) approaches the operational wavelength  $\lambda$ . The form of the mode pattern in single-mode fibers is well described by a Gaussian function of the form

$$\psi(x',y') = \exp\left[-\left(\frac{r'}{r_0}\right)^2\right]$$
(14.69)

The Gaussian mode is completely specified by the radius  $r_0$  at which the amplitude drops to its  $1/e^2$  value. Recalling Eq. 14.57, the mode profile at the fiber end also governs the  $1/e^2$  far-field divergence angle

$$\theta = \tan^{-1}\left(\frac{\lambda}{\pi w_0}\right) \approx \frac{\lambda}{\pi w_0}$$

if  $w_0 = r_0$  is the waist radius of the mode profile at the  $1/e^2$  intensity.

#### 14.4.2 Multi-Mode Fibers

As their name implies, multi-mode fibers propagate more than one mode. The number of modes depends on the core radius a and numerical aperture (NA) and is given by  $V^2/2$ , with

$$V = \frac{2\pi}{\lambda_0} a \sqrt{n_1^2 - n_2^2} = \frac{2\pi}{\lambda_0} a n_1 \sqrt{2\Delta}$$
(14.70)

V is known as the *normalized frequency* or *waveguide parameter*. As the value of V increases, the number of modes supported by the fiber increases. A step-index fiber becomes single-mode for a given wavelength when V < 2.405.

Three parameters are required to specify a step-index or graded-index multi-mode fiber: the refractive index of the core material  $n_1$ , the refractive index of the cladding material  $n_2$  and the radius of the cylindrical core a.

The mode pattern of the fundamental mode in a weakly guiding fiber is given by

$$\psi(r') = \begin{cases} \frac{A}{J_l(U)} J_l\left(\frac{Ur}{a}\right) \left[\frac{\cos l\phi}{\sin l\phi}\right], & r < a \\ \frac{A}{K_l(W)} K_l\left(\frac{Wr}{a}\right) \left[\frac{\cos l\phi}{\sin l\phi}\right], & r > a \end{cases}$$
(14.71)

where

$$U = a \left(k_0^2 n_1^2 - \beta^2\right)^{1/2}$$
(14.72)

$$W = a \left(\beta^2 - k_0^2 n_2^2\right)^{1/2}$$
(14.73)

 $k_0 = 2\pi/\lambda$  and  $\beta$  is known as the propagation constant and  $r = \sqrt{x^2 + y^2}$ . For guided modes we must have  $k_0^2 n_2^2 < \beta^2 < k_0^2 n_1^2$ , or with the normalized propagation constant

$$b = \frac{\beta^2 / k_0^2 - n_2^2}{n_1^2 - n_2^2} = \frac{W^2}{V^2}$$
(14.74)

we must have 0 < b < 1. We can then write the eigenvalue equations for the mode structure

$$V(1-b)^{\frac{1}{2}} \frac{J_{l-1}\left(V(1-b)^{\frac{1}{2}}\right)}{J_{l}\left(V(1-b)^{\frac{1}{2}}\right)} = -Vb^{\frac{1}{2}} \frac{K_{l-1}\left(V(b)^{\frac{1}{2}}\right)}{K_{l}\left(V(b)^{\frac{1}{2}}\right)}, \qquad l \ge 1$$

$$V(1-b)^{\frac{1}{2}} \frac{J_{1}\left(V(1-b)^{\frac{1}{2}}\right)}{J_{0}\left(V(1-b)^{\frac{1}{2}}\right)} = -Vb^{\frac{1}{2}} \frac{K_{1}\left(V(b)^{\frac{1}{2}}\right)}{K_{0}\left(V(b)^{\frac{1}{2}}\right)}, \qquad l = 0$$
(14.75)

where J, K are the J- and K-Bessel functions. For a given value of l, there will be a finite number of solutions of the eigenvalue equations (Eq. 14.75) and the  $m^{th}$  solution (m = 1,2,3,...) is referred to as the  $LP_{lm}$  mode.

A derivation of this mode structure can be found in Gloge [15] and Ghatak [13]. The maximum number of modes N is approximated by

$$N \approx \frac{V^2}{2} \tag{14.76}$$

for V >> 1.

OpTaliX calculates the mode structure for all possible modes in a multi-mode fiber and performs a coupling efficiency calculation for each mode separately. The individual results are combined for a total coupling efficiency.

Note that computing time will increase significantly with increasing number of modes calculated on both source and receiver fiber, because CEF must be computed for each mode combination separately. For example, allowing only 10 modes in both source-fiber and receiver-fiber results in 100 separate calculations of coupling efficiency. It is therefore recommended to limit the maximum number of *calculated* modes by the FSMM and FRMM commands.

#### 14.4.3 Display Fiber Modes

The individual modes of a multi-mode fiber can be displayed using the MMF command, which opens a dialog box for editing fiber parameters (see Fig. 14.33).

Compute modes for a step i	index fiber		spiritoris
Fiber Parameter	-	Copy field to	()
Core Index Cladding Index Core Radius	1.510000 1.500000 0.02500	Bitmap INT-File	
LM-Mode LM=14	<b>•</b>	Close Dialog	

Figure 14.33: Calculation and display of fiber modes.

The maximum number of modes that can be calculated and displayed is 200. Fiber parameters such as core index, cladding index and core radius can be explicitly specified in the appropriate fields or obtained from predefined fibers from the pull-down menu. Note that on selecting new fiber parameters, the program automatically searches for all possible modes (¿ 200), which may take a while depending on the parameters selected and on computer speed. Clicking on the "Compute Mode Field" button displays the selected mode profile. The intensity of the mode field can be saved as bitmap file (BMP, PNG or PCX) or INT-file (Code V compatible).

#### 14.4.4 Fiber Coupling Example 1

As our first example, we choose a SELFOC<sup>TM</sup> SLW10 gradient index rod-lens from NSG and for source and receiving fiber a single-mode fiber SMF28 from Corning is selected. This configuration, as shown in Fig. 14.34 on the next page, can be found in the examples library (selfoc-coupler.otx). The pitch of the gradient index lens has been adjusted to 0.5, which gives unit magnification and therefore optimum coupling conditions for the selected fibers.



Figure 14.34: Coupling of two Corning SMF28 fibers with NSG-SELFOC<sup>TM</sup> lens SLW10.

From the main menu, selecting *Diffraction Analysis*—— >*Fiber Coupling*, invokes a dialog box (Fig. 14.35), which allows editing of all relevant coupling parameters. In this example, they are already preselected from the fiber catalogue. Mode-field radius and  $1/e^2$  divergence are automatically updated, if a fiber is selected from the catalogue. The source fiber is assumed at the selected field position (as defined by the XOB and YOB commands) and the receiving fiber is assumed at the position of the chief ray coordinates in the image plane.

**Important:** The correct amplitude distribution in the pupil of the coupling optics is automatically calculated by the transformation process from the source fiber end to the entrance pupil. It is therefore not necessary to adjust the amplitude profile by the apodization parameter PUI, PUX and PUY. In order to obtain correct results in fiber-to-fiber coupling, PUI, PUX and PUY shall be 1. Check the corresponding settings.

Only in the special case of a parallel laser beam entering the coupling optics (object at infinity) should the apodization be properly adjusted, since transformation of the source will be skipped for this condition.

📢 Fiber Coupling Efficiency	
Source (Fiber or Diode)	Receiving Fiber
Mode Profile © Gaussian © Fundamental step-index	Mode Profile © Gaussian © Fundamental step-index
X         Y           1/e^2 radius         0.00521         0.00521           Far field divergence         0.09494         0.09494           Core index         1.510000           Cladding index         1.50000           Core radius         0.02500           Tilt around X-axis         0.000           Tilt around Y-axis         0.000           Other parameter         Size of FFT grid :           1         1	1/e^2 radius       0.00521       mm         Far field divergence       0.09494         Core index       1.510000         Cladding index       1.50000         Core radius       0.02500         Tilt around X-axis       0.000         Tilt around Y-axis       0.0000         X-displacement       0.0000         Y-displacement       0.0000         Fix fiber location in image plane at
Cancel	X = 0.00000 Y = 0.00000
	Help

Figure 14.35: Dialog box showing coupling options for the setup shown in Fig. 14.34.

```
Fiber Coupling Efficiency:
Field number
                     : 1
                                   0.0000/
                                              0.0000)
                              (
Image coordinates
                                   0.0000/
                                             0.0000)
                     :
                              (
                     : 1
Wavelength number
                                   1.5500 micron )
                              (
Transformation grid
                     : 64
                            SOURCE
                                          RECEIVER
                                                    Unit
Fiber type
                     :
                           SMF-28
                                           SMF-28
1/e^2 radius
                                          0.00520
                          0.00520
                     :
                                                      mm
Far-field divergence :
                         0.09488
                                          0.09488
                                                     rad
Tilt around X-axis :
                                          0.00000
                          0.00000
                                                     dea
Tilt around Y-axis
                     :
                           0.00000
                                           0.00000
                                                     deg
X-displacement
                                           0.00000
                                                      mm
                     :
Y-displacement
                                           0.00000
                     :
                                                      mm
Transmission
                     : not considered
                          0.99271 ( -0.032 dB)
Power coupling
                  :
                          0.99953 ( -0.002 dB)
Power coupling (ideal):
```

This example shows very little basic insertion loss (-0.032dB), since the NA of the coupling optics is about 2.1 times larger than the fiber divergence (0.09488). The ideal power coupling (-0.002dB) is the theoretical maximum efficiency if the optics introduced no aberrations and does not truncate the beam. It is a representation how good source fiber and receiving fiber match.

#### 14.4.5 Fiber Coupling Example 2

The second example will be a demultiplexer, which we load from the examples library (demux.otx). Since the design employs a diffraction grating, it is basically a spectrometer, which separates the wavelengths (channels) into different fibers.



Figure 14.36: A simple demultiplexer, shown at only one wavelength.

The system is defined at three wavelengths, which describes the spectral range of interest. We will also switch to "spectrometer" mode (this relates all aberrations to the current wavelength, rather than to the base wavelength), which is currently only possible from the configuration dialog (from the main menu, select *Edit*— ->*Configuration* and then the tab "General").

We will now define a user defined graphics UGR (see section 12.10, page 206) to plot coupling efficiency (CEF) versus wavelength. User defined graphics is found under the *tools menu*. In the dialog to appear, predefined settings may be restored. We will do so and restore (load) from the macro subdirectory cef\_vs\_wl.ugr. All settings should be right for our example and we immediately run the plot.



Figure 14.37: Coupling efficiency versus wavelength.

# **Illumination Analysis**

The illumination option is used to compute the illuminance/radiance distribution at any surface of the system, including the image surface. As opposed to point-like objects (defined by "fields", see sect. 7.3.1, page 44), illumination sources are extended in the spatial domain. OpTaliX currently supports two types of illumination sources,

- **flat emitting sources**. There are predefined flat sources, such as circular, elliptical or rectangular flat shapes, Gaussian, double pinhole, or flat sources defined by bitmap images.
- **ray sources**, that is, sources defined by a collection of rays.

**Point sources** (fields) are defined in the *optical system configuration* (see sect. 7.3.1, page 44) and are *always* located on the object surface. Thus, object coordinates ("fields") are always referred to the vertex of the object surface. The location of the object surface itself is defined, for example, by the object distance (S0), x-decenter of the object surface (XDE s0), etc.

**Sources used in illumination calculations** *always* exhibit a finite spatial extension and their locations may be referred either to the global coordinate system or the object coordinate system. See page 29 for definition of coordinate systems.

#### **15.1** Commands for Defining Illumination Sources

Command line entries for illumination source parameters allow two forms: a long form and a short form. Note that the short form is required in defining zoom/multi-configuration systems.

Also, do not confuse the qualifier "sk" used for sources and surfaces. In this section, and for illumination purposes only, "sk" is exclusively used for sources. For all other commands, not related to illumination or source properties, "sk" always refers to surfaces!

	Allocates memory for N_max sources and defines the up-
	per limit of allowable sources. MAXSRC is only required if
	more than 200 illumination sources (the default value) are
MAXSRC N_max	required.
	This command must not be confused with the subsequent
	command SRC, which defines the number of actually used
	sources used in an optical system.
	continued on next page

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SRC n_sources	Without any other qualifier SRC n_sources specifies the number of sources used in the optical model. Example: src 3 ! specifies 3 sources.	
SRC sk TYPE [FIL file_name] Short form: Sxxx sk	Example: src 3 ! specifies 3 sources. Defines source type. The command exists in a long and short form. sk is the source number. The short form i required in zoom definitions and LDM queries. In the lon, form, TYPE can be any one of CIR top hat circular ELL top hat elliptical REC top hat rectangular GAU Gaussian BMP Bitmap file (*.BMP, *.PCX, *.PNG) INT INT file GRA Grating PIN Double pinhole CHE Checker board RAY Rays defined in file_name In the short form, xxx is a place holder for the source type It is defined as follows: SCIR top hat circular SELL top hat elliptical SREC top hat rectangular SGAU Gaussian BMP Bitmap file (*.BMP, *.PCX, *.PNG) SINT INT file SGRA Grating SPIN Double pinhole SCHE Checker board Examples: src s1 ELL ! top hat elliptical source, srec s2 ! short form: top hat rectangular source no.2, src s2 RAY FIL c:\rayset.dat ! ray source.	
SRC USE sk Y N Short form: SUSE sk Y N	Use source sk. Once defined, sources can be in- cluded or excluded in illumination ray trace. The short form is required in zoom definitions and LDM queries. Examples: src s1 use y ! Source 1 is used (included) in illumination analysis, src s2 use n ! source 2 is ignored (excluded) in illumination analysis.	

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	Source sk is referenced to object coordinate system (O) or global coordinate system (G).	
SPC DEE at OLC	Examples:	
Short form: SCREE sk OLC	src s1 ref o ! Source 1 is referred to object	
Short Ionn. Server Sk 0 9	coordinate system,	
	sgref s2 g ! source 2 is referred to global co-	
	Source total emitted power.	
SRC PWR sk power	Examples:	
	source 1 is 1.0 Watts	
Short form: SPWR sk power	source 1 is 1.0 watts.	
	3 Watts.	
SRC sk XEXT x_ext		
Short form: SXEX sk x_ext	Defines source X-extension (in mm). sk is the source num-	
	ber. If omitted, sk defaults to source 1. See also Fig. 15.6.	
SRC sk YEXT y_ext		
Short form: SYEX sk x_ext	Defines source Y-extension (in mm). sk is the source num-	
	ber. If omitted, $sk$ defaults to source 1. See also Fig. 15.6.	
SRC XDE sk x_dec		
Short form: SXDE sk x_ext	Defines source X-decenter (in mm). Decenter is measured	
	from the vertex of the source coordinate system (object or	
	to source 1. See also sect. 15.2 for definition of source	
	coordinate system.	
SRC YDE sk y_dec		
Short form: SYDE sk y_dec	Defines source Y-decenter (in mm). Decenter is measured	
-	from the vertex of the source coordinate system (object or	
	global). sk is the source number. If omitted, sk defaults	
	to source 1. See also sect. 15.2 for definition of source	
	coordinate system.	
SRC ZDE sk z_dec		
Short form: SZDE sk z_dec	Defines source Z-decenter (in mm). Decenter is measured	
	from the vertex of the source coordinate system (object or global), giving the source number. If omitted, giving defaults	
	to source 1 See also sect 15.2 for definition of source	
	coordinate system.	
SRC ADE sk x_tlt		
Short form: SADE sk x_tlt	Tilt of source normal about X-axis (in degrees). sk is the	
	source number. If omitted, sk defaults to source 1. See	
	also sect. 15.2 for definition of source coordinate system.	
SRC BDE sk y_tlt		
Short form: SBDE sk v_tlt	Tilt of source normal about Y-axis (in degrees) sk is the	
	source number. If omitted, sk defaults to source 1. See	
	also sect. 15.2 for definition of source coordinate system.	
	continued on next page	

continued from previous page	
SRC CDE sk z_tlt	
Short form: SCDE sk z_tlt	Tilt of source normal about Z-axis (in degrees). sk is the source number. If omitted, sk defaults to source 1. See also sect. 15.2 for definition of source coordinate system.
SRC DIVX sk div_x	
Short form: SDIVX sk div_x	X-divergence of source emission (in degrees), full with. sk is the source number. If omitted, sk defaults to source 1.
SRC DIVY sk div_y	
Short form: SDIVY sk div_y	Y-divergence of source emission (in degrees), full with. sk is the source number. If omitted, sk defaults to source 1.
SRC AOFFS sk	
ang_offset_alpha	
Short form: SOFA sk ang_offset_alpha	Angular offset $\alpha$ of source emission from the source normal (in degrees) in the Y/Z plane. See also Fig. 15.2. sk is the source number. If omitted, sk defaults to source 1.
SRC BOFFS sk	
ang_offset_beta	
Short form: SOFB sk ang_offset_beta	Angular offset $\beta$ of source emission from the source normal (in degrees) in the X/Z plane. See also Fig. 15.2. sk is the source number. If omitted, sk defaults to source 1.
SRC COS sk	
cos_power_factor	
Short form: SCOS sk cos_power_factor	Cosine power factor. Defines source emittance as a function of the emittance angle. sk is the source number. If omitted, sk defaults to source
	The intensity of rays emitted from an extended source can be controlled by the cosine power factor (SCOS) in
	dependence of the angle at which the ray is launched from the source normal. The emitted ray intensity is described by the following function:
	$I_{ray} = \cos(\alpha)^{SCOS} \tag{15.1}$
	where $\alpha$ is the angle at which the ray is emitted and SCOS is the cosine power factor. See also section 15.3.1 for a more detailed description.
	Examples:
	SCOS $0.0$ : All rays are emitted at the same inten- sity, irrespective of the emittance angle at which the ray is launched.
	SCOS 1.0 : Ray intensity follows the Lambertian Law, $I = cos(\alpha)^{1.0}$
	continued on next page

continued from previous page	
SRC ARAY sk analysis_rays	
Short form: SARAY sk analysis_rays	Source analysis rays. Number of rays traced in illumina- tion analysis for source sk. If sk is omitted, source 1 is assumed.
SRC PRAY sk plot_rays	
Short form: SPRAY sk plot_rays	Source plot rays. Number of rays displayed in layout plots for source sk.
SRC WAV sk	
source_wavelength_number	
Short form:	Source wavelength number. $0 = $ all wavelength.
SWAV sk wavel_number	
LIS SRC [sk]	List illumination sources. sk is the source number. If sk is absent, all sources defined are listed.
ILL SAV Y N	Save illumination data along with prescription data, Y=yes, N=no.

## **15.2 Illumination Sources Coordinate Definition**

The position and orientation of flat and real sources may be freely chosen in 3D space. As described in 15.3 sources may be referred to the object coordinate system or the global reference coordinate system (see also the SGREF command). If the illumination source is referred to the object surface, its position and orientation also depend on the object surface location/orientation. Fig. 15.1 shows the dependencies of source position and orientation with respect to the object surface.

## **15.3 Defining Illumination Sources in the GUI**

Source parameters can also be defined in dialogs from the graphical user interface (GUI). From the command line, invoke the illumination dialog by

ILL [?]       Runs illumination analysis. The optional parameter "?" invokes a di alog box for editing illumination parameter prior to illumination anal ysis.
----------------------------------------------------------------------------------------------------------------------------------------------------------------

or from the main menu *Geom.Analysis* -> *Illumination*. Because illumination sources are mostly extended objects, in contrast to the point-like objects normally used in optical analysis (also called 'field objects'), illumination (extended) sources may also defined in the configuration dialog. It is invoked by

EDI CNF	Edit configuration parameters. Select the Illum.Source tab to define
	illumination source parameters.

The following graphic (Fig. 15.3) shows the dialog for defining various illumination sources.



Figure 15.1: Definition of source coordinate system in relation to object coordinate system.

#### 15.3.1 Controlling Source Emittance Characteristics

The emittance characteristics of a source, i.e. its apparent intensity as a function of the viewing angle from the source normal, can be defined for flat sources (circle, rectangle, etc.) by the SCOS parameter. The emitted intensity as a function of the emittance angle  $\alpha$  is described by

$$I(\alpha) = I_0 \cdot \cos(\alpha)^{SCOS} \tag{15.2}$$

Figure 15.4 indicates the effect of the SCOS parameter on the angular emittance function.

Note that the SCOS parameter is ineffective for sources that are defined by a collection of rays ("ray sources").

#### 15.3.2 Controlling Source Rays in the Lens Layout Plot

An important means to control the correct setting of source parameters is the visualization of rays emitted by the sources. By default, plotting of rays emanating from (extended) sources is disabled in the layout plot. Because analysis of illumination sources usually involves a massive amount of rays, this would significantly slow down rendering of sources (and the rays) in the lens layout plot. Source rays, however, can be enabled in lens layout plots by enabling the check box "*Show illumination source rays*" in the option dialog box (right click in the lens layout window), as shown in Fig. 15.5



Figure 15.2: Angular offsets (SOFA, SOFB in degree) of source emission relative to source normal.

#### **15.3.3** Flat emitting Sources

The illumination option allows specification of flat sources, such as circular, elliptical or rectangular flat shapes, Gaussian, double pinhole, etc. Flat sources are defined on a plane surface only, as indicated in Figure 15.6. Flat sources emit at a constant intensity at every point of the source area confined by (SXEX, SYEX).

Note that standard field specifications, as defined for point sources in the "fields" tab of the optical system configuration (EDI CNF), are ignored in illumination analysis.

Wavelength weights (WTW) are used to model the spectral transmission of the system, not the source. Initially, all sources are emitting spectrally uniformly at all specified wavelengths. Wavelength weights will then act as a spectral filter applied to the source.

A flat source (object) is defined by its full extension in X- and Y-direction (SXEX, SYEX). The source is located at (SXDE, SYDE, SZDE) with respect to the reference system which is either the global coordinate system or the object coordinate system. The flat surface may also be tilted by the angles (SADE, SBDE, SCDE) to indicate an emission direction different from the coordinate Z-axis.

The light emission is confined in a cone defined by the divergence parameters (SDIVX, SDIVY).

#### **15.3.4** Flat Source with Gaussian Profile

Flat sources with a Gaussian profile are characterized by a non-uniform intensity across the source area. The profile is scaled to the source extensions SXEX, SYEX, such that the 50% of the peak intensity is obtained exactly at 1/3 of the source extension, the 1/e2 intensity is obtained at 0.567 of the source extension, and the source intensity at the rim of the source extension is 0.1954%. Fig. 15.7 illustrates these relationships.

#### **15.3.5** Sources defined by Rays

A volume source models any real-world source such as an incandescent lamp, LED, or laser diode. Instead of defining a precise geometrical model, the radiant source is modelled in OpTaliX by a three-dimensional space-angular source characterization in terms of a collection of rays, in the following called *ray source*.

Additional parameter are enabled or greyed out depending on source type. 🕯 Illumi General Source Target Plot Style Define type and placement of light sources. This can be a flat emitting object (circle, rectangle, etc), a source image stored as a bitmap or INT-file, or a source defined by ray. Number of sources : 2 🗧 Use Source type Source file Browse Ref. XEXT YEXT Rays DivX AngOffs X Enable or disable Top hat rectangula 1.000 1.0000 50.00 50.00 0.00 Dbject source in illumination 1.0000 1.0000 1000 30.00 30.00 0.00 Top hat rectangular Object analysis Select source type (circular, elliptical, rectangular, from bitmap, etc) F Help Cancel OK Calculate File name containing ray data Source is referred to object (only for ray sources). or global coordinate system

Figure 15.3: Dialog for defining illumination sources. Invoked by commands ILL ? or by EDI CNF.

Individual rays in a "ray source file" are defined by spatial ray coordinates (X, Y, Z), direction cosine  $(\alpha, \beta, \gamma)$ , intensity and wavelength, stored in a user supplied file. Rays provided in a "ray source file" must obey to the file format as given in sect. 32.13.

Ray sets (i.e. a collection of rays) defining a source may also be generated from third party software provided by other vendors, such as

- ASAP: These are ray files in a binary format originally defined and mainly used in the optical analysis package ASAP. The typical extension of these files is '\*.dis',
- IES TM-25 is an industry standard of a uniform data format for ray files. The extension is '\*.TM25RAY',
- ASCII: Ray sets are defined in a text file using the standard ASCII character coding. The file format is explained in section 32.13, page 525.

Rays emanating from a source are assumed to be located either at the object coordinate system or the global coordinate system. Sect. 5.2 (page 29) describes these coordinate systems.

#### 15.3.6 Source Rays aimed to System Entrance Pupil

In some cases it might be difficult to trace a sufficient number of rays emitted from an illumination source through the optical system. In the wide-angle system, as illustrated in Fig. 15.9, the majority of the emitted rays are wasted because they don't pass through the narrow entrance aperture. One would normally increase the number of source rays in order to obtain a decent number of rays at the target (image) surface.

In order to avoid this inefficient situation, a second option is offered by which rays from the extended source are directly aimed to the entrance pupil, instead of blindly launched from the source within the



Figure 15.4: Effect of SCOS parameter on the angular emittance of a source, shown in a polar diagram.

specified emittance cone. In the illumination ray aiming option, the source emittance characteristics is then completely ignored. Fig. 15.10 indicates the definition of illumination rays for this option.

Note that this option requires dedicated selection on how the source itself and the entrance pupil are sampled. For example (compare with Fig. 15.10),

Object sampling = 50: Divides the source area in 50 x 50 cells from which source rays are randomly generated.

Pupil sampling = 8: From each object cell, 8 x 8 rays are aimed to the entrance pupil.

In total, 50x50x8x8 = 160000 rays are then used for each particular source and wavelength.

#### 15.3.7 Ray Source Viewer

"*Ray sources*" are sources defined by a collection of rays. The ray data is stored in plain ASCII files. Even though the data may be viewed in conventional ASCII editors, typically the sheer amount of data prevents a thorough understanding and interpretation of the source itself. The "*ray source viewer*" option provides a means for visualizing this data.

In addition to only viewing ray data, ray sets may also be transformed (shifted, rotated) and subsequently saved as a new ray file.

The ray source viewer is invoked from the command line by

VIE SRC FIL source_file	View ray source defined in source_file. The file name of the ray source may have extensions *.txt, *.dat, or *.ray for plain ASCII formats, respec- tively *.dis for the ASAP binary format. Other ray formats will be added later.
-------------------------	-------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------

or from the main menu: Display - Ray Source Viewer. A dialog box is invoked which allows viewing orientation (azimuth, elevation), zoom, and visualization of arrows indicating the ray direction.

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📢 LensDraw	
Plot Surface Range 🛛 📮 to 🛛 7 🚔	Plot Options
	Draw Surface Number
Plot Wavelengths :	Enable edge plotting
Plot Scale : 5.0000	Show Aperture Bounds
(0=automatic)	Check Heights
Perspective View Plot Offsets	Suppress Frame
Azimuth 90.00 × 0.0000	Auto-update Rays
Elevation 21.00 Y 0.0000	Asymmetric Apertures (AAP)
z 0.0000	Hide dummy surfaces
	Show surface operdinate system
Page Format 🛛 🗛 Landscape 💌	Show illumination source rays
	Plot Rays
	<ul> <li>Default</li> </ul>
	Fan, X/Z-Plane
	C Fan, Y/Z-Plane
Cancel OK	C Fan, X/Z- and Y/Z-Plane
	O Fan, aperture circumference

Figure 15.5: Enabling plot of source rays in lens layout plot. The setting is saved with the lens prescription.

Figure 15.12 shows the source represented by ray coordinates and ray directions proportional to the ray intensity.

#### 15.3.8 Transforming Ray Data

Source rays may be arbitrarily transformed in 3D-space. This is accomplished from within the ray source viewer dialog (see previous section).

Note that applying a transformation is cumulative. In order to 'undo' a transformation you must apply shift/rotate parameters with reverse sign. If more that one transformation (e.g. shift + rotation) is simultaneously applied and if you want to undo (reverse) this operation, you should keep in mind that coordinate transformations are not commutative (i.e. depend on order of operation). From this point of view it is advisable to apply only one parameter at a time. The result of ray transformation is then immediately visible in the ray source viewer.

Once transformed, ray data may also be stored in a separate file for later use. Select a file name and export the transformed ray data by pressing the Export button in the dialog shown above (Fig. 15.13). Two different output formats are provided, ASCII or binary. Note that the binary file format for OpTaliX ray sources is compatible to the ASAP binary format.

#### **15.4** Illumination Analysis Options

ILL [?]	Runs illumination analysis. The question mark invokes a dialog box for setting of parameters prior to analysis.
	continued on next page

continued from previous page		
ILL SAV Y N	Store illumination data with prescription data, Y=yes, N=no.	
ILL EXP FIL out_file [RAW INT XLS]	Save irradiance distribution at target surface to file. Re- quires preceding illumination analysis (use ILL com- mand above). The full path specification including file extension must be given. The specific file format is rec- ognized by one of the file extensions, RAW (raw file, ASCII-format), TXT (raw file, ASCII-format), INT (in- terferogram file) or XLS (Excel file). The default file format option is RAW.	
ILL TAR sk	Target surface for illumination. This is the surface at which the irradiance distribution is computed. Examples: ill tar s5 ! Illumination target surface is 5, ill tar si ! Illumination target surface is image sur- face.	
ILL IMX x_ext	X-image extension (full width) of analysis region at target surface.	
ILL IMY y_ext	Y-image extension (full width) of analysis region at target surface.	
ILL NXI X_Img_Cells	Divides the image (target) extension IMX into NXI cells.	
ILL NYI Y_Img_Cells	Divides the image (target) extension IMY into NYI cells.	
ILL FIL out_file [RAW INT XLS]	Save irradiance distribution at target surface to file. The full path specification must be given. The specific file format is defined by one of the (optional) parameters, RAW (raw file), INT (interferogram file) or XLS (Excel file). The default file format option is RAW.	
RPWR	Database item: Return total received power, including all activated sources, using illumination ray tracing. Ex- ample: eva [rpwr]	
EPWR	Database item: Return emitted power from all activated sources. Example: eva [epwr]	
NILR	Database item: Return number of successfully received illumination rays at target surface, including all active sources. Example: eva [nilr]	



Figure 15.6: Definition of flat (surface-like) sources.



Figure 15.7: Definition of a Gaussian source. The profile is scaled to the source extensions SXEX, SYEX.



Figure 15.8: Coordinate system for defining rays in a "ray-source" model.



Figure 15.9: Aiming source rays to entrance pupil.

v <sup>4</sup> Illumination	X
General Source Target Plot Style	
Zoom positions       1       to       1         Low level       0.001000       Relative measure. ( 0.01 = 1% )         Calculation Method       •       Launch rays from source as defined (preferred)         •       Use ray aiming to entrance pupil (ignore source emittance characteristics)         Object sampling       20       Pupil sampling         8       •	
Help Cancel OK Calculate	

Figure 15.10: Selecting alternative illumination option: Aiming source rays to the entrance pupil directly. The number of rays traced per source is  $(objectsampling)^2 \cdot (pupilsampling)^2 \cdot NumberOfColours$ 



Figure 15.11: Dialog for visualizing ray source data.

Figure 15.12: Visualization of ray data. Left: Shows ray coordinates only (arrow length = 0), right: Arrow length  $\geq 0$ . The length of the arrows indicates relative intensity of the rays.

📢 Ray Source		
View Transform/Export		
Coordinate transformation of ray data. Rays origi and rotated. Transformed ray data may then be transformations (shift and rotate) are cumulative. apply it with opposite sign.	nating from a source may be arbitrarily shifted exported (written) to a file. Note that In order to undo a transform operation you must	
Shift Source Source X-Decenter 0.00000 Source Y-Decenter 0.00000 Source Z-Decenter 0.00000	Rotate Source       Rotation about X-Axis       Rotation about Y-Axis       90.00000       Rotation about Z-Axis       0.000000	Step 1: Enter transformation data.
Export transformed ray data to file:		Step 2: Apply transformation.
	Browse	
Export every 1 🚼 ray Power 17.675	Export	
Help	Close	

Figure 15.13: Transformation (shift, rotate) of ray data.

## **16**

## **Physical Optics Propagation**

#### (Diffraction Based Beam Propagation)

Optical modelling consists largely of geometrical ray tracing in which the light is represented by a set of rays which are normal to the wavefront. Diffraction effects in "conventional" systems, such as a photographic objective, are small and localized to the edge of the beam. Rays are used to determine the pupil function and do a far-field diffraction analysis. This is a fast and well established method to calculate diffraction PSF and MTF, as described in sections 14.2.1 and 14.2.2.

This method, however, breaks down if noticeable diffraction occurs inside optical systems. A common example is a simple spatial filter (pinhole) located at the focal point of a laser system. Ray optics is unable to predict removal of the phase aberrations by the pinhole. Also, it cannot account for the beam spreading of Gaussian beams. In this context, note that the Gaussian beam analysis (BEA) as described in section 14.3 only models *paraxial* quantities of ideal Gaussian bemas and does not include wave aberrations.

For such cases, physical optics methods must be used. It models a *coherent* optical beam by a complex-valued function (amplitude and phase), describing the transverse beam distribution. In the computer, the beam is represented by a complex 2-dimensional array of discretely sampled points. The entire array (beam) is then propagated through the optical system. This approach is also commonly called *diffraction based beam propagation*.

Physical optics propagation is based on several algorithms, which are described in the following sections. For a detailed study of the underlying physical principles, see Goodman [17].

#### 16.1 Propagation of the Angular Spectrum

If the complex field (amplitude and phase) is Fourier-transformed across any plane, the various spatial Fourier components can be considered as plane waves travelling in different directions. The field across any other plane can be calculated from the phase shifts these plane waves have undergone during propagation.

Let us assume a wave field  $U(x, y, z_1)$  incident on a plane and we wish to obtain the resulting field  $U(x, y, z_2)$  across a second, parallel plane at distance z to the right of the first plane. At the z = 0 plane the two-dimensional Fourier transform ( $\mathcal{F}$ ) of the field U is given by

$$A(f_x, f_y, 0) = \iint_{-\infty}^{\infty} U(x, y, z_1) e^{-2\pi j (f_x x + f_y y)} dx dy$$
(16.1)

and correspondingly U can be obtained from the inverse Fourier transform  $(\mathcal{F}^{-1})$  of its spectrum,

$$U(x, y, z_1) = \iint_{-\infty}^{\infty} A(f_x, f_y, z_1) e^{2\pi j (f_x x + f_y y)} df_x df_y$$
(16.2)

Physically the integrand of Eq. 16.2 can be interpreted as a plane wave propagating with wave vector  $\vec{k}$  with magnitude  $2\pi/\lambda$ . It has direction cosines  $(\alpha, \beta, \gamma)$  as shown in Fig. .... The complex phasor amplitude of the plane wave across a constant z-plane is given by

$$P(x, y, z) = e^{j\overrightarrow{k}\overrightarrow{r}} = e^{\frac{2\pi j}{\lambda}(\alpha x + \beta x)}$$
(16.3)

The complex exponential function  $e^{2\pi j(f_x x + f_y y)}$  may be regarded as representing a plane wave propagating with direction cosines

$$\alpha = \lambda f_x \tag{16.4}$$

$$\beta = \lambda f_y \tag{16.5}$$

$$\gamma = \sqrt{1 - (\lambda f_x)^2 - (\lambda f_y)^2}$$
 (16.6)

The complex amplitude of the plane wave component is evaluated in the Fourier domain of U at the spatial frequencies  $f_x = \alpha/\lambda$ ,  $f_y = \beta/\lambda$ . Hence, the function

$$A(f_x, f_y, z_1) = \iint_{-\infty}^{\infty} U(x, y, z_1) e^{-2\pi j (f_x x + f_y y)} dx dy$$
(16.7)

is called the angular spectrum of the field  $U(x, y, z_1)$ . The angular spectrum of U across a plane parallel to the  $z_1$  plane but at a distance z from it is written in the form

$$A(f_x, f_y, z_2) = A(f_x, f_y, z_1) exp\left[\frac{2\pi j}{\lambda} \Delta z \sqrt{1 - (\lambda f_x)^2 - (\lambda f_y)^2}\right]$$
(16.8)

Thus, propagation of a complex field from one plane to another can be written in terms of operators for Fourier transform  $\mathcal{F}{U(z_1)}$  and free space propagation  $\mathcal{T}{z_2 - z_1}$ 

$$U(z_2) = \mathcal{F}^{-1} \left[ \mathcal{T} \{ z_2 - z_1 \} \mathcal{F} \{ U(z_1) \} \right]$$
(16.9)

This is a straightforward procedure in which the input field is Fourier transformed (i.e. decomposed into its frequency components), the plane wave propagator applied (i.e. adding the relative phases of the components of the angular spectrum) and then the resulting distribution inverse Fourier transformed. Since the angular spectrum method can only propagate a field between parallel planes, we will subsequently refer to it as the plane-to-plane (PTP) operator.

The direction cosines of the plane waves must satisfy the condition

$$\alpha^2 + \beta^2 < 1 \tag{16.10}$$

otherwise evanescent waves are obtained, which are not covered by the angular spectrum model.

#### **16.2** Propagation using the Fresnel Approximation

In the Fresnel approximation the field  $U(x, y, z_2)$  is calculated from the initial field  $U(\xi, \eta, z_1)$  where the propagation distance is  $\Delta z = z_2 - z_1$ . The field is given by

$$U(x, y, z_2) = \frac{e^{jkz_2}}{j\lambda\Delta z} e^{\frac{jk}{2\Delta z}(x^2 + y^2)} \iint_{-\infty}^{\infty} \left\{ U(\xi, \eta, z_1) e^{\frac{jk}{2\Delta z}(\xi^2 + \eta^2)} \right\} e^{-j\frac{2\pi}{\lambda\Delta z}(\xi x + \eta y)} d\xi d\eta \qquad (16.11)$$

This is the Fourier transform of the complex field at the initial plane multiplied by a quadratic phase exponential. It can also be written in operand notation

$$U(z_2) = \left[\frac{e^{jkz_2}}{j\lambda\Delta z}\right] \mathcal{Q}\{x, y, \Delta z\} \mathcal{F}\left[\mathcal{Q}\{\xi, \eta, \Delta z\} U(\xi, \eta, z_1)\right]$$
(16.12)

where  $\mathcal{Q}{\xi, \eta, \Delta z} = e^{\frac{jkr^2}{2\Delta z}}$  is the quadratic phase exponential with  $r^2 = \xi^2 + \eta^2$ . The term  $\mathcal{Q}{\}$  outside the integral may be omitted if the resultant field is referred to a sphere of radius z instead a plane. At this point it is worthwhile to remember that the field is actually defined on a parabola (quadratic approximation), however, within the scope of the Fresnel approximation we have already assumed  $(\xi, \eta) << z$ . Referring the phase to a sphere is the preferred choice, since the phase variations are much smaller rather than referring the field to a plane. Eq. 16.12 can now be redefined as the waist-to-sphere (WTS) operator

$$U(z_2) = \left[\frac{e^{jkz_2}}{j\lambda\Delta z}\right] \mathcal{F}^s\left[\mathcal{Q}\{\xi,\eta,\Delta z\}U(\xi,\eta,z_1)\right]$$
(16.13)

and

$$s = \frac{\Delta z}{|\Delta z|} \tag{16.14}$$

The sphere-to-waist (STW) propagation is obtained by reversing the operations,

$$U(z_2) = \left[\frac{e^{jkz_2}}{j\lambda\Delta z}\right] \mathcal{Q}\{x, y, \Delta z\} \mathcal{F}^s \left[U(\xi, \eta, z_1)\right]$$
(16.15)

Note that the term  $e^{jkz_2}$  in equations 16.13 and 16.15 can normally be neglected, since it is a constant phase propagation term.

Using a Fast Fourier Transform (FFT) algorithm and representing the field in a two-dimensional complex-valued array, the sampling period at the  $z_2$  plane or sphere is not constant but scales linearly by

$$\Delta x = \frac{\lambda |\Delta z|}{N \Delta \xi} \tag{16.16}$$

where N is the number of sampling points in the array.
# **16.3** Propagation through Optical Interfaces

The angular spectrum and Fresnel propagators are used for propagating through homogeneous space. At optical interfaces the complex transmittance function of optical elements (lenses, diffractive surfaces, aspheres, etc) are required to calculate the complex field after the element. Since these functions are not analytically known (except in the strict paraxial approximation), a combination of classical ray tracing and wave optics is used. This requires conversion of the field after free space propagation into rays, doing refraction/reflection at the optical interface and converting the resultant rays back into the complex field description.

#### 16.3.1 Converting Field into Rays

The field is assumed at a sphere or plane, which is the result from a previous propagation operator (angular spectrum or Fresnel). The complex wave amplitude at the coordinates (x, y) in a two-dimensional array of data points is given by

$$U(x_m, y_n) = a(x_m, y_n)e^{j\Phi(x_m, y_n)}$$
(16.17)

where a is the amplitude and  $\Phi$  is the phase in  $2\pi/\lambda$  units. The coordinates  $(x_m, y_m)$  are assumed to form an equidistant mesh. Since the wave-optical propagation delivers the phase modulo  $2\pi$ , a phase unwrapping algorithm must be used. This is, in the absence of noise, a straightforward operation. Following an arbitrary continuous path through the gridded data, the following decision rule is applied:

$$\Phi_{k+1} = \begin{cases} \Phi_k + \Delta_k - 2\pi & \text{if } \Delta_k > \pi \\ \Phi_k + \delta_k + 2\pi & \text{if } \Delta_k < \pi \\ \Phi_k + \delta_k & \text{else} \end{cases}$$
(16.18)

where k is the path index and  $\Delta_k$  is is the adjacent-pixel phase difference. From the unwrapped phase the ray direction vector  $\vec{v}$  is obtained by

$$\overrightarrow{v} = \frac{\lambda}{2\pi} \left[ \frac{\partial \Phi}{\partial x}, \frac{\partial \Phi}{\partial y}, \sqrt{\left(\frac{\lambda}{2\pi}\right)^2 - \left(\frac{\partial \Phi}{\partial x}\right)^2 - \left(\frac{\partial \Phi}{\partial y}\right)^2} \right]$$
(16.19)

#### 16.3.2 Transfer at Optical Interfaces

Starting from the input reference sphere, the ray is traced through the optical interface to the output reference sphere using geometric optics techniques. See also Fig. 16.1. Generally, input sphere and output sphere will be in the immediate vicinity of the optical interface.

The phase  $\Phi$  is derived from the path length L of the ray between input reference and output reference and is added to the complex input field.

$$L = \frac{2\pi}{\lambda} \sum n_i \cdot L_i \tag{16.20}$$

where  $n_i$  is the index of refraction along the sub-path  $L_i$ . The total optical path may include a single optical interface or even a series of interfaces (surfaces).



Figure 16.1: Relationship between diffraction-based beam propagation and geometrical ray tracing shown at the example of a Gaussian beam.

#### 16.3.3 Converting Rays into Field

The phase  $\Delta \Phi$  introduced in the geometric ray trace section of the path is derived from the optical path length between input sphere and output sphere and is added to the phase component of the complex field. Real and imaginary parts of the output field are then obtained by

$$R = a(x_m, y_n)\cos(\Phi + \Delta\Phi)$$
(16.21)

$$I = a(x_m, y_n)\sin(\Phi + \Delta\Phi)$$
(16.22)

If the output mesh is substantially distorted, resampling of the data points into a rectangular grid must be performed.

# **16.4** Propagation Control

Surrogate Gaussian beams are used to determine the algorithms to be used. These beams are considered to represent approximately the actual beam and since they have an easily calculated width at all points in space, they allow a convenient method of determining the size of the two-dimensional array holding the field data. Any complex input field may be approximately fit to a Gaussian beam of radius  $\omega$  and phase radius R. From these values, the Gaussian waist size  $\omega_0$  and the distance to the waist  $z_w$  are calculated. The radius  $R_1$  of the input sphere is then obtained by

$$R_1(z) = z \left[ 1 + \left( \frac{\pi \omega^2}{\lambda z} \right) \right]$$
(16.23)

where z is the distance from the waist. The radius  $R_2$  is calculated by the lens law

$$\frac{1}{R_1} - \frac{1}{R_2} = \frac{1}{f} \tag{16.24}$$

where f is the focal length of the optical interface. Since the beam spreads due to diffraction it may overfill the array. Fortunately, near-field propagators (angular spectrum) and far-field propagators

(Fresnel) may be combined to control the size of the array so that aliasing due to the finite sampling is sufficiently suppressed. The sampling period of the near-field (angular spectrum) propagator is constant, while the sampling period of the far-field (fresnel) propagator scales linearly with propagation distance  $\Delta z$  according to Eq. 16.16. An appropriate transition point from a constant sampling period to a linearly scaling sampling period is chosen by the Rayleigh range  $z_R = \omega_o^2 \pi / \lambda$ . This choice minimizes the phase error if a plane reference inside the Rayleigh distance and a spherical reference outside the Rayleigh distance is selected. Fig. 16.2 indicates the array sizes inside and outside the Rayleigh range.

The control of the propagation algorithm should allow movement from any point in space to any other. To do so the previously defined primitive operators, plane-to-plane (PTP), waist-to-sphere (WTS) and sphere-to-waist (STW) are appropriately combined. We define four new operators, which cover all possible cases (see also Fig. 16.2)

$$\mathbf{II}(z1, z2) = \mathbf{PTP}(z_2 - z_1)$$
 inside  $z_R$  to inside  $z_R$   

$$\mathbf{IO}(z1, z2) = \mathbf{WTS}(z_2 - z_{\omega})\mathbf{PTP}(z_{\omega} - z_1)$$
 inside  $z_R$  to outside  $z_R$   

$$\mathbf{OI}(z1, z2) = \mathbf{PTP}(z_2 - z_{\omega})\mathbf{STW}(z_{\omega} - z_1)$$
 outside  $z_R$  to inside  $z_R$   

$$\mathbf{OO}(z1, z2) = \mathbf{WTS}(z_2 - z_{\omega})\mathbf{STW}(z_{\omega} - z_1)$$
 outside  $z_R$  to outside  $z_R$   

$$\mathbf{OO}(z1, z2) = \mathbf{WTS}(z_2 - z_{\omega})\mathbf{STW}(z_{\omega} - z_1)$$
 outside  $z_R$  to outside  $z_R$   

$$\mathbf{OO}(z1, z2) = \mathbf{WTS}(z_2 - z_{\omega})\mathbf{STW}(z_{\omega} - z_1)$$
 outside  $z_R$  to outside  $z_R$   

$$\mathbf{OO}(z1, z2) = \mathbf{WTS}(z_2 - z_{\omega})\mathbf{STW}(z_{\omega} - z_1)$$
 outside  $z_R$  to outside  $z_R$ 

The primitive operators are defined in equations 16.9, 16.13 and 16.15 respectively.



Figure 16.2: Variation of array size inside and outside the Rayleigh range. The four different possibilities in propagating inside/outside the Rayleigh range are indicated by the acronyms II, IO, OI, OO.

For practical usage of the algorithms described above, three major issues should be considered:

- The sampling interval,
- the oversizing of the array relative to the beam size,
- and the use of reference surfaces.

The sample spacing  $\Delta x$  and  $\Delta y$  determines the highest spatial frequency, which can be represented. The region of space which is covered by the whole array is  $M\Delta x$  and  $N\Delta y$ , where M, N are the number of sample points in x- and y-direction. The sample spacing and the array size should be chosen as to overfill the beam by a factor 3-5. The choice of this factor depends largely on the profile of the input beam. For Gaussian profiles a factor 3 may be appropriate while for top hat functions factors of 5-10 are recommended. If the width of the array is too small, aliasing will occur. Aliasing is due to the discrete sampling and the finite extent of the computer arrays. Because of propagation a collimated beam expands and the field may grow beyond the array bounds. The portions of the beam which fall outside the array then "fold back" and will cause aliasing.

# **16.5 Command Overview**

EDI BPR	
	Invokes a dialog box for editing beam propagation parameter. Currently, param-
	eters can only be defined in the dialog, there are no equivalent commands yet.
	See a detailed description of the relevant parameters in the following section 16.6
	(Propagation Parameters).
BPR	
	Executes beam propagation and displays resulting field.

# **16.6 Propagation Parameters**

📢 Physical Optics Propagation (POP)	(S <sup>SL</sup> PI	ysical Opt	ics Propag	ation (POP)					×
Beam Definition Propagators	Bea	Definition	Propagator	rs					
Sampling 256 V Wavel 1 Grid oversize factor 5 Input Field 1 on surface 1 Object width X 1.00000 Object width Y 1.00000	0E 51 2 3 4	Propaga PTP PTP PTP	ator 1 Fix	Propagator 2 PTP PTP PTP PTP V	Fix	21 0.000 -20.000 -40.000 -100.000	22 20.000 40.000 100.000 0.000	Rayleigh         ▲           7068.583         7068.583           7068.583         785.398           785.398         785.398	[
Graing Period     0.04000       File     Browse       Output Field     File       on surface     5       Compute Fiber Coupling Integral     Plot Phase (20)       Plot Phase (20)     Plot Phase (cross sections)									
Help Calculate Cancel OK			Help	Calculate		Cancel	ОК		<u> </u>

Figure 16.3: Parameter dialogs of the free-space propagation example.

The first tab of the dialog (see Fig. 16.3), labelled 'Beam Definition', defines the parameter of the beam and other auxiliary propagation parameter.

#### **Beam Definition Tab:**

- **Sampling:** Defines the number of sampling points across the data grid. This number is somewhat arbitrary, however, it should be noted that accuracy of simulation increases with higher numbers. Low numbers ( $\leq 128$ ) should only be selected if there is little high spatial frequency content in the source profile (such as Gaussian) and if little spreading of the beam is expected. 'Top-hat' profiles contain relatively high spatial frequency components (due to the sharp edge) and therefore sampling numbers  $\geq 256$  should be selected. Also note that computing time goes with the square of the sampling number, that is computing time is 4 times higher on 256 sampling points as compared to a 128 sampling.
- **Grid oversize factor:** Defines the physical size of the array in relation to the beam dimensions. The array must always be larger as to overfill the beam by the grid oversize factor and ensures that all frequency components of the beam profile are contained in the array. This factor also depends on the beam profile. Typical values are 3-5 for Gaussian beams, 8-10 for 'top-hat' profiles.
  - **Object type:** Select from several predefined profiles. (Import from a file not yet functional).
  - **Object width:** Specifies the maximum physical extension of the source beam in X-direction and Y-direction respectively. The physical extension of the array used in beam propagation is then 'grid oversize factor' \* max(object\_width\_X, object\_width\_Y).
- **Input field surface:** The surface number where the source beam (object) is placed and where from the propagation starts.
  - **Grating period:** This field is only accessible for amplitude grating sources and defines the grating period (one cycle) in X-direction.
- **Output field surface:** The surface number at which the propagation is terminated and the field components are displayed.
- Fiber Coupling Integral: Takes the resultant field and convolves it with the profile of a receiving fiber in order to compute coupling efficiency.

#### **Propagators Tab:**

#### **Propagator:** There are 5 types of propagators:

PTP: Plane-to-Plane. Uses the angular spectrum method (sect. 16.1) to propagate a field from a plane surface over a distance z to another plane surface.

WTS: Waist-to-Sphere. Propagates a field defined on a plane surface (near the beam waist) over a distance z to a spherical (reference) surface, using the Fresnel approximation (sect. 16.2). The distance z must be 2 times larger than the Rayleigh range.

STW: Sphere-to-Waist. Propagates a field defined on a spherical surface (far from the beam waist) over a distance z to a plane (reference) surface, using the Fresnel approximation (sect. 16.2). The distance z must be 2 times larger than the Rayleigh range.

Ray: Does a conventional ray trace (ignores diffraction) over the distance z. This propagator is used in GRIN media (where FFT propagation fails) or where diffraction effects are expected to be neglected. This speeds up calculation.

Blank: A blank field means, no propagation is performed.

**Fix:** If checked, fixes (freezes) propagator selection and overrides automatic propagator selection. See also notes below.

#### Notes:

The program traces a pilot ray through the optical system. This is a paraxial Gaussian beam and allows very rapid finding of the location of waists with respect to surfaces, calculation of Rayleigh range and calculation of the reference spheres/planes at the optical surfaces. On this basis, the best propagator is selected and displayed in the dialog box (see Fig. 16.3, right). This selection can be overruled by the user by checking the appropriate check boxes in the columns 'Fix 1' and 'Fix 2' respectively.

Propagation between surfaces is typically performed in two steps, using two propagators successively. To illustrate the point, consider Fig. 16.4

Since there is no Sphere-to-Sphere propagator (yet), the field is first propagated from the reference sphere at surface 2 to the waist location over the distance  $z_1$ , using a STW (sphere-to-waist) propagator. From this location the field is propagated to the reference sphere at surface 3 over the distance  $z_2$  (in negative direction).

This is why two propagators are offered for each surface in the BPR dialog (Fig. 16.3). The Rayleigh range  $z_R$  is a convenient measure for selecting the appropriate propagator.

$$z_R = \omega_o^2 \pi / \lambda \tag{16.26}$$

where  $\omega_o$  is the beam radius (semi-diameter). The Rayleigh range indicates that axial range around the waist where the field (the wavefront) may still be considered with good accuracy as plano. Outside the Rayleigh range, beam spreading and wavefront curvature are noticeable. We also refer to the operators description in Eq. 16.25 and Fig. 16.2 to describe the four possible cases of propagation.

The simplest case is the 'inside-inside' (II) case. That is, propagation distance z is less than the Rayleigh range  $(-z_R \text{ to } + z_R)$ . The radius of the wavefront is infinity or nearly infinity. Thus, a beam



Figure 16.4: Propagation from surface 2 to 3.

travelling inside this range may be well modelled by the angular spectrum method, which propagates between plano (infinity radius of curvature) surfaces. Therefore, this propagator is called **PTP** (plane-to-plane).

If the propagation distance is larger than the Rayleigh range  $z_R$ , the **IO** case ('inside-outside'), respectively the **OI** case ('outside-inside') apply. The radius of the wavefront at the start surface (OI case) respectively at the receiving surface (IO case) is no longer infinity. The Fresnel approximation is now used as propagator, which propagates a field from a sphere to a waist (STW) respectively from a waist to a sphere (WTS).

# 16.7 Examples

The examples to follow give a step-by-step introduction to propagating coherent (monochromatic) beams through optical systems. All the OpTaliX files referred to in the subsequent sections are found in the examples directory optalix examples pop

# **16.7.1** Free-Space Propagation

Fig. 16.5 shows the optical setup for propagating a plane wave over a certain distance in free space. The predefined OpTaliX file is found under \optalix\examples\pop\freespace.otx. The input field is a 'top-hat' amplitude profile defined by a circular screen (aperture) of 1mm diameter on surface 1. We will calculate the field at the subsequent surfaces 2-5, which are placed at various distances to the screen (surface 1).

1 2 3 4

Figure 16.5: Optical setup for simple free-space propagation

The BPR dialog (click on the BPR icon underneath the main menu or enter EDI BPR in the command line) shows suitable predefined parameter for this example: The beam starts at surface 1 with a diameter of 1mm and a circular 'top-hat' amplitude profile. Since the we start with a plane wave the waist is also at surface 1. The size of the grid array is  $256 \times 256$  and it overfills the beam by a factor 5.

The output surface, i.e. the surface on which the output field is displayed may be freely selected between 1 and 5. The resulting fields are shown in Fig. xxx.

Figure 16.6: Fields at various propagation distances.

#### 16.7.2 Talbot Imaging

The Talbot imaging phenomenon is present for any periodic structure. At a specific distance, defined by the wavelength and the period of the periodic structure (typically an amplitude grating), a perfect image is obtained. A multiplicity of such images appear behind the grating, without the help of lenses. The z-locations at which the perfect image (also called a self-image) can be observed must satisfy the condition

$$z = \frac{2nL^2}{\lambda} \tag{16.27}$$

where L is the period of the periodic structure and n is an integer.



Figure 16.7: Talbot imaging

Note that the side lobes are due to the finite extent of the grating structure.

# 16.7.3 Coupling Efficiency Example

This example uses a symmetrical optical configuration to couple the output of a single mode fiber into another single mode fiber. The design file is found under

\optalix\examples\pop\coupling-efficiency.otx. We have seen in section 14.4 (page 294) that fiber coupling efficiency (CEF) algorithms based on geometrical ray tracing predict coupling efficiency reasonably well if diffraction effects inside the optical system can be neglected.

We will now consider a case where diffraction effect play a significant role. The axial separation between the aspheric coupling lenses is 200mm. Due to the small diameter the beam will spread out (diverge) as it propagates in the free space. Due to diffraction, the beam diameter at the receiving lens will be larger than predicted by purely geometric ray tracing and the wavefront will no longer be plano. That gives rise to a different location of the focus position as compared to the geometric spot.



Figure 16.8: Fiber coupling 1:1 relay optics.

The source and receiving fibers are standard Corning SMF-28 types with  $5.2\mu m$  mode field radius. Since the fibers are single mode, their emitted respectively exited field is close to a Gaussian and we may run a Gaussian beam analysis (see BEA option in sect. 14.3) in order to obtain a first quick overview about the expected the beam parameters:

an Beam Analy	sis:					
ength = ared =	1.55000 micron 1.00000					
lane :						
Spot Size	Waist Size	Waist Dist	Divergence	RFR Radius	Rayleigh R	. Fresnel
SRY	WRY	ZWY	GDY	RCY	RRY	No.
0.005200	0.005200	0.00000	0.094598		:	Inf
0.005200	0.005200	0.00000	0.065612	-0.14440E+21	0.054806	0.003
0.338163	0.294006	99.561456	0.001678	0.40786E+03	175.198763	0.738
0.294007	0.294006	-0.438544	0.001678	-0.69992E+05	175.198763	0.558
0.338893	0.005189	5.146211	0.065750	0.51474E+01	0.054574	14.399
0.005189	0.005189	0.000146	0.094797	0.20344E+02	0.054574	1000000.000
0.005189	0.005189	0.000146	0.094797	0.20344E+02	0.054574	
	an Beam Analy ength = ared = lane : Spot Size SRY 0.005200 0.338163 0.294007 0.338893 0.005189 0.005189	an Beam Analysis: ength = 1.55000 micron ared = 1.00000 lane: Spot Size Waist Size SRY WRY 0.005200 0.005200 0.005200 0.005200 0.338163 0.294006 0.294007 0.294006 0.338893 0.005189 0.005189 0.005189	an Beam Analysis: ength = 1.55000 micron ared = 1.00000 lane: Spot Size Waist Size Waist Dist SRY WRY ZWY 0.005200 0.005200 0.000000 0.005200 0.005200 0.000000 0.338163 0.294006 99.561456 0.294007 0.294006 -0.438544 0.338893 0.005189 5.146211 0.005189 0.005189 0.000146 0.005189 0.005189 0.000146	an Beam Analysis: ength = 1.55000 micron ared = 1.00000 lane: Spot Size Waist Size Waist Dist Divergence SRY WRY ZWY GDY 0.005200 0.005200 0.000000 0.094598 0.005200 0.005200 0.000000 0.065612 0.338163 0.294006 99.561456 0.001678 0.294007 0.294006 -0.438544 0.001678 0.338893 0.005189 5.146211 0.065750 0.005189 0.005189 0.000146 0.094797 0.005189 0.005189 0.000146 0.094797	an Beam Analysis: ength = 1.55000 micron ared = 1.00000 lane: Spot Size Waist Size Waist Dist Divergence RFR Radius SRY WRY ZWY GDY RCY 0.005200 0.005200 0.000000 0.094598 0.005200 0.005200 0.000000 0.065612 -0.14440E+21 0.338163 0.294006 99.561456 0.001678 0.40786E+03 0.294007 0.294006 -0.438544 0.001678 -0.69992E+05 0.338893 0.005189 5.146211 0.065750 0.51474E+01 0.005189 0.005189 0.000146 0.094797 0.20344E+02 0.005189 0.005189 0.000146 0.094797 0.20344E+02	an Beam Analysis: ength = 1.55000 micron ared = 1.00000 lane: Spot Size Waist Size Waist Dist Divergence RFR Radius Rayleigh R SRY WRY ZWY GDY RCY RRY 0.005200 0.005200 0.000000 0.094598 0.005200 0.005200 0.000000 0.065612 -0.14440E+21 0.054806 0.338163 0.294006 99.561456 0.001678 0.40786E+03 175.198763 0.294007 0.294006 -0.438544 0.001678 -0.69992E+05 175.198763 0.338893 0.005189 5.146211 0.065750 0.51474E+01 0.054574 0.005189 0.005189 0.000146 0.094797 0.20344E+02 0.054574 0.005189 0.005189 0.000146 0.094797 0.20344E+02 0.054574

We see that the focus, i.e. the location of the waist, is practically identical to the position of surface 6. The geometric analysis (use spot or fan aberration plots), however, indicates a clear defocus.

This example is also a good exercise for selecting the correct propagators based on the Rayleigh range. For example, propagation from surface 2 to 3 over 100mm distance is completely within the Rayleigh range ( $z_R = 175.199mm$ ), so the PTP operator will be initially proposed by the program. The waist, however, is not exactly at surface 3 but 0.439mm in front of surface 3. Since propagation is always performed from and to the waist, the program proposes propagation in two steps, first PTP over 99.561mm and secondly PTP over 0.439mm. Since surface 3 is so close to the waist, we override the program's choice by disabling the second propagator. Check the 'Fix' check box and select a blank field in the menu. That will also reduce computation time. In a future release, the program will automatically recognize such conditions.

In order to calculate coupled energy, the receiving fiber must be specified. Click on the 'Fiber Parameter' button in the 'Output Field' section of the dialog. A new dialog will be opened. In fact, this is the

📢 Physical Optics Propagation (POP)	📢 Phy	sical Optics Pr	opag	ation (POP)			_
Beam Definition Propagators	 Beam	Definition Prop	agator	s			
Samples 129 - Manual 1		Propagator 1	Fix	Propagator 2	Fix z1	z2	Rayleigh 🖄
Sampling 120 V Waver.	OBJ	<b></b>	•	<b>v</b>	0.000	0.000	0.055
Grid oversize factor 10 🗧 Field 1	1	<u> </u>	2	wts 🔽	0.000	5.146	0.055
	STO	PTP 🔻	•	- I-	99.561	0.439	175.199
Input Field:	3	<u> </u>	~	PTP 🔻	-0.439	100.439	175.199
on surface 1 Object width X 0.01040	4	STW 💌	~	PTP 🔽	5.146	0.000	0.055
Dhiect width Y 0.01040	5	<u> </u>	~	- L-	0.000	0.000	0.055
Ubject type CORNING SMF-28  Grating Reside 0.02000							
citating Period   0.02000							
File Browse							
Output Field							
on surface 5							
Plot field (cross sections)							
Compute Fiber Coupling Integral Plot Phase (2D)							
Fiber Parameter Plot Phase (cross sections)							
							-
	1						
Help Calculate Cancel OK		Help	1	Calculate	Cancel	OK	
			_				

Figure 16.9: Dialogs for physical optics based calculation of coupling efficiency

dialog used in the CEF option (geometrical ray trace based) where only the receiving fiber parameters may be edited. The source fiber (source field) parameters are greyed out because the source field is already specified in the BPR dialog.

The output in the text window is:

BEAM PROPAGATION : Source Parameter: Object width : X = 0.01040 Y = 0.01040 Object patch : X = 0.10400 Y = 0.10400 Sampling : 128 Source type : CORNING SMF-28 Linear coupling efficiency : 0.9935 Coupling loss : -0.0283 dB

As already expected from the Gaussian beam analysis (BEA) shown on page 332, coupling is nearly perfect. In contrast to this result, the geometric optics based CEF option calculates a relatively high loss, which corresponds to the defocus of the geometric spot.

```
Linear coupling efficiency : 0.619749
Coupling loss : -2.0778 dB
```

# 16.8 Restrictions

Diffraction beam propagation assumes *coherent* (monochromatic) radiation. Partial coherence or non-monochromatic light cannot be modelled by this option.

In the current implementation, only axial conditions can be modelled. Decentered and/or tilted configurations or skew beams should be avoided. This capability is subject to later releases.

# 17

# **Transmission Analysis**

Computes the transmittance of a single ray or a bundle of rays through the optical system. The transmission is computed as a fraction of the incident intensity which is normalized to 1 (i.e. 100%). The transmission calculation accounts for vignetting due to clipping apertures or obscurations, ray losses (clipping due to ray trace errors), reflection losses at coated or uncoated surfaces, material bulk absorption, gaussian pupil apodization, surface intensity filters and the polarization state of the source radiation.

Calculation of the transmittance can be controlled in OpTaliX by four options (see also Fig. 17.1).

- 1. Absorption of radiation *within* optical materials is controlled by the TRA command. Use TRA yes or TRA no to activate/deactivate bulk material transmittance in calculations.
- 2. Reflection losses at optical interfaces (coated or uncoated) are controlled by the POL command, which activates/deactivates polarization ray tracing. See POL yes | no command to include/exclude effects from coated or uncoated surfaces.
- 3. Intensity filters (surface apodization) modify the intensity transmission along a ray path. These filters may be loaded from INT-files and associated to optical surfaces.
- 4. The system pupil may be apodized using the commands PUI, PUX, PUY. This feature is mainly used to model non-uniform source radiation such as lasers.



Figure 17.1: Effects on transmission.

Thus, in order to calculate transmission through an optical system including the effects of bulk material absorption and surface reflection losses, the following options must be activated:

TRA yes POL yes

Likewise, the combination TRA yes, POL no, includes the effects of material absorption but ignores all surface reflection losses, whether they are coated or not.

If polarization ray trace is enabled (POL yes), output of transmission analysis depends on the polarization state of the source radiation. Use the POLSTATE command to select between polarized or unpolarized input radiation (see also section 18, page 343). By default, the source radiation is assumed unpolarized.

Bulk absorption losses of each material in the optical system are obtained from the glass types. Absorption losses are dependent on the integrated path-length, the material and the wavelength. If bulk absorbtion data is not available for a given glass (e.g. for fictitious glasses), the transmission along the ray path in this material will be assumed 100%.

# 17.1 Effect of Coatings/Cement on Transmission

By default, each air-glass surface is assumed to be uncoated, i.e. the Fresnel reflections at each air/glass interface are computed, if polarization ray trace is activated (POL yes). Mirrors without coating specification are assumed as "perfect" (100%) reflectors.

Attach real multilayer coatings to surfaces (see also ATT command on page 389) in order to get most accurate results. Multilayer coatings may be loaded, analyzed and optimized in the coatings menu and then assigned (attached) to any surface. The surface can be converted to an uncoated surface using the DEL MUL command.

A default coating can be applied on each surface for transmission analysis. It is assumed to be single layer  $MgF_2$  with a quarter wave thickness normal to the surface at the reference wavelength. The default coating is defined and attached to a surface by the

#### ATT si..j|k DEF

command (see also ATT command on page 389), or by entering DEFCOAT in the coating column of the surface editor. An example is shown in Fig. 17.2

													De on	efines a sing surfaces 1	gle N - 2	MgF <sub>2</sub>	layer
<b>\(<sup>®</sup> Su</b>	rface Edi	tor: E:\optalix\ex	am	ples\Misc\DOU	BLE	_GAUSS.OTX										_	
Stand	lard Data	Decenter, Tilts A	sphe	ere GRIN Sol	ves	Special Aperture	s	Hologram 🛛	Mis	2.							
	TYPE	Radius		Distance		GLASS		APE-Y	×.	Shape	GIb	THR		Comment		loating	
OBJ	S	0.0000000		0.1000000E+21			_	0.00	0	circular 💽		0.00000				5	
1	S	28.7248827		4.373329		BSM24		15.00	1	circular 💽		0.00000		(	DEF	COAT	
2	S	94.2300334		0.1490908				14.60	0	circular 🔄		0.00000			DEF	COAT	/-/
3	S	17.4436362		6.212115		SK1		12.71	0	circular 🔄		0.00000					
4	S	0.0000000		1.888483		F15		12.26	0	circular 🔄		0.00000					
5	S	10.7346033		7.553932				8.48	0	circular 🔄		0.00000					
4																	
EFL = MAG	FL = 50.00024 BFL = 31.56893 EPD = 25.00000 ₩ PIM MAG = 0.000000 SYL = 37.52117 0AL = 69.04452																
Pos.	1 🔻	Insert Surf. Inse	rt File	e Delete Surf.		Help Clos	e										

Figure 17.2: Defining a "default" coating (single MgF2 layer) on surfaces.

Cemented surfaces (glass-glass interfaces) are assumed uncoated; the transmission losses are derived from Fresnel reflection losses caused by the index difference of the two adjacent materials. In order to exactly model the effect of cement, split the cemented surface into two surfaces which enclose the cement material.

# 17.2 Transmission along Chief Ray

By default, transmission is based on the chief ray tracing only. Thus, only one ray (the chief ray) is used to calculate transmission. Using this option, all aperture related effects are ignored. In particular for systems with large numerical apertures, large field angles or large ray incidence angles at surfaces, transmission analysis which integrates over the aperture should be preferred (see section 17.3).

**Command syntax:** 

TRA yes no	Includes bulk absorption in transmission analysis. "Yes", includes bulk absorption effects in all subsequent calculations (e.g. PSF, MTF).
	"No" ignores transmission effects and the aperture is assumed uni-
	formly illuminated (except when apodization of the system has been
	explicitly specified, see commands PUI,PUX,PUY.
TRA STEPS n_steps	Number of wavelength intervals (steps) within the wavelength range
	below).
TRA LAM [FIL	Plot (chief ray) transmission vs. wavelength (LAM). Transmission data
filename]	may be exported to a file (in ASCII or Excel format) if a file name
	following the FIL qualifier is specified. Note that the extension of
	the file specification determines the file format (.txt or .dat for
	ASCII format, .x1s for Excel format).
TRA FLD	Plot (chief ray) transmission vs. field
TRA SUR	Plot chief ray transmission decomposed to surface contributions at
	all fields and wavelengths. For aperture averaged analysis add the
	optional parameter AVG to this command (section 17.3).
TRA NUM	Print chief ray transmission for all fields and wavelengths defined in
	the optical system. See also transmission integrated over the aperture
	in section 17.3).
	Mean Transmission along a single ray. Only available as lens
	database item (LDI). Example:
	eva [tra si f1 w3 z4 0 1]
TRA fk wk sk zk	Calculates transmission at surface si (image) along single ray de-
	fined at field 1, wavelength number 3, zoom position 4. The data
	pair (0 1) defines the relative coordinates in the entrance aperture.
	The example here describes the marginal Y-ray in the pupil.
	Transmission for S-polarized light along a single ray. Only avail-
	able as lens database item (LDI). Example:
	eva [tras si fl w3 z4 0 1]
TRAS fk wk sk zk	Calculates S-pol transmission at surface si (image) along single
	ray defined at field 1, wavelength number 3, zoom position 4.
	The data pair (01) defines the relative coordinates in the entrance
	aperture. The example here describes the marginal 1-ray in the
	pupil. Transmission for S-polarized light along a single ray. Only avail-
	able as lens database item (I DI). Example:
	eva [trap si f1 $w$ 3 74 0 1]
	Calculates P-pol transmission at surface si (image) along single
TRAP fk wk sk zk	ray defined at field 1 wavelength number 3 zoom position 4
	The data pair (0.1) defines the relative coordinates in the entrance
	aperture. The example here describes the marginal Y-ray in the
	pupil.
TRR	Print transmission of user defined plot rays. See the commands SET
	RAY and SET FAN in section 190 for definition of various ray bun-
	dles.

#### Example:

We assume a simple achromatic doublet and attach the standard 3-layer coating "ar\_1" (W-type antireflection coating) from the coating library to surfaces 1 and 2. We leave surfaces 3 and 4 uncoated.

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This is accomplished by the commands, assuming the doublet is already in use:

att s1..2 file ar\_1 ! Attach coating "ar\_1" to surfaces 1 - 2 tra sur ! compute transmission vs. surfaces

The incident intensity is always 1. The output gives the relative intensity along the chief ray. As shown below, transmission values are listed at each wavelength. The ratio of output to input intensity is given for each source of loss, where reflection losses are designated REF and absorption losses (occurring in the bulk material) are designated ABS.

Wav	rel.:	0.400	0.450	0.500	0.550	0.600	0.650
	Fie	eld 1					
REF:	0	1.0000	1.0000	1.0000	1.0000	1.0000	1.0000
REF: ABS: REF:	1 2	0.9747 0.9980 0.9747	0.9990 0.9990 0.9990	0.9982 0.9990 0.9982	0.9968 0.9990 0.9968	0.9991 0.9990 0.9991	0.9996 0.9990 0.9996
REF: ABS: REF:	3 4	0.9085 0.9697 0.9085	0.9124 0.9960 0.9124	0.9149 0.9988 0.9149	0.9166 0.9994 0.9166	0.9179 0.9994 0.9179	0.9188 0.9994 0.9188
Total		0.7588	0.8268	0.8322	0.8336	0.8397	0.8422

This example shows the effects of surface reflection losses and bulk absorption losses. Since no coating is specified at surfaces 3 and 4, Fresnel reflection losses are calculated for these surfaces. Fresnel reflection R on *uncoated* surfaces for normal incidence is given by

$$R = \left(\frac{n-1}{n+1}\right)^2 \tag{17.1}$$

Note also the steep falloff of transmission at shorter wavelengths (400-450nm), which is caused by bulk absorption in the second lens and the lower antireflection efficiency of this coating in the blue spectrum.

# **17.3** Transmission integrated over Aperture

A bundle of rays is traced through the optical system which fills the entire pupil. The output of this analysis is the mean transmission value of all rays. Note that this calculation is computing intensive and the result may be outputted delayed, depending on computer speed. The transmission calculation accounts for vignetting due to clipping apertures or obscurations, ray losses (clipping due to ray trace errors), losses at coated and uncoated surfaces and material bulk absorption.

TRA LAM AVG	Plot transmission vs. wavelength (LAM), integrated over full aperture.
TRA FLD AVG	Plot transmission vs. field, integrated over full aperture.
TRA SUR AVG	Plot and list transmission integrated over full aperture and decom-
	posed to surface contributions at all fields and wavelengths.
TRA NUM AVG	Print transmission integrated over aperture for all fields and wave-
	lengths defined in the optical system.

#### **Command syntax:**

A sample output for the 'TRA NUM AVG' command is shown below:

```
TRANSMISSION ANALYSIS (full aperture):
TRA yes
POL no
Wavelength: 0.656 0.588 0.486
----- Field 1 ------
Transmittance :
                          0.9626 0.9787
                                                       0.9803
Proj. solid Angle 0.1937 0.1939
                                                      0.1938

        Effective NA
        0.2483
        0.2484

        Relative Illum.
        1.0000
        1.0000

                                                        0.2483
                                                         1.0000
 ----- Field 2 ------
Transmittance :0.96270.9787Proj. solid Angle0.14180.1419Effective NA0.21240.2125
                                                         0.9805
                                                        0.1405

        Effective NA
        0.2124
        0.2125

        Relative Illum.
        0.7321
        0.7319

                                                        0.2115
                                                         0.7252
 ----- Field 3 ------
Transmittance : 0.9637 0.9793
                                                        0.9809
Proj. solid Angle 0.0966 0.0962 0.0956

        Effective NA
        0.1753
        0.1750

        Relative Illum.
        0.4991
        0.4964

                                                      0.1745
                                                        0.4939
```

For each field, wavelength and zoom position, output reports transmittance, projected solid angle, effective numerical aperture and relative irradiance.

- Transmittance includes losses at air-glass interfaces (coated or uncoated surfaces) and material absorption losses. Set POL yes to enable air-glass losses and TRA yes to enable absorption losses.
- Proj. solid Angle Defines the solid angle of the bundle of rays as seen from the image point. This is purely a geometric factor and corresponds to the square of the apparent numerical aperture  $(sin(u)^2)$  at a given field. Vignetting (i.e. truncation of the beam) decreases this value.
  - Effective NA Related to the projected solid angle and describes the effective numerical aperture at a given field.
  - Relative Illum. The product of transmittance and projected solid angle. A graphical representation of this value is obtained by the RIRR command (relative irradiance, see following section). The relative irradiance is dimensionless and is always referred to the first field.

# **17.4 Relative Irradiance**

RIRR [NUM]	Plots relative irradiance at the image surface. Includes field depen-
	dent cosine effects and vignetting. Set POL yes to include air-glass
	losses and TRA yes to include material absorption losses. The op-
	tional parameter NUM outputs numerical data.

Plots the relative irradiance (also called relative illumination) in image space by determining the apparent size of the exit pupil in direction cosine space, including all effects like distortion, vignetting, pupil aberration, wavelength weighting and system transmission. The size of the exit pupil is calculated by tracing a bundle of rays through the optical system which fills the entire entrance pupil. NRD (number of rays across diameter) controls accuracy of the result as well as speed of calculation. The higher NRD, the more accurate the result will be, however, computation time increases quadratically with NRD.

The relative irradiance is the apparent off-axis pupil area divided by the pupil area of the first field defined in the system. Note that the apparent pupil area in OpTaliX is expressed by the solid angle (in sin(u) units) as seen from the image point. This approach is valid for any general optical system and not limited to rotationally symmetric systems. A detailed treatment of calculating relative illumination is found in [42].

Use POL yes and TRA yes to include transmission losses on air-glass interfaces (including coatings) and losses due to bulk absorption.

#### Note:

If the system is badly aberrated, the solid angle calculations obtained from ray trace may no longer provide accurate results for relative irradiance. In this case, accurate results are obtained by reversing the system with the image surface modelled as the object surface. Then the product of the transmittance and the projected solid angle in object space gives the relative irradiance with high accuracy, regardless of aberrations.

# **17.5** Colour Contribution Index

The colour code describes the influence of photographic lenses on the colour rendition of colour films. It is applicable only to the visible wavelength range, i.e. between approximately 370nm and 680nm and is only defined on-axis. Although the colour code is only defined at the optical axis, OpTaliX calculates a colour code for all given fields, indicating possible colour shifts as a function of the field. This feature is particularly interesting in wide angle applications. This calculation also takes into account the effects of multilayer coatings, if attached to surfaces (see also section 20 and how to attach coatings to optical surfaces).

The colour contribution index is calculated according to the following scheme (ISO 6728) :

Compute the spectral (wavelength-dependent) transmission  $T(\lambda)$  in 10nm intervals in the range 370 - 680nm. The spectral transmission is then multiplied with the spectral sensitivity (weight)  $W(\lambda)$  of a standard photographic film, as given in the following equation and in table 17.1 :

$$T_{eff} = \sum T(\lambda) \cdot W(\lambda) \tag{17.2}$$

The total photographic responses,  $R_B$ ,  $R_G$ ,  $R_R$ , are expressed as  $Log_{10}$  values, i.e.

$$R_B = \log_{10} \left( T_{eff\_blue} \right) \tag{17.3}$$

Likewise,  $R_G$  and  $R_R$  are determined. Finally, the smallest element of this three number designation is equaled to zero by subtracting it from all three log values.

#### **Command syntax:**

CCI	[AVG]	[fij	zij]	Calculates the colour contribution index (CCI) according
				ISO 6728 (1983) for each field and zoom position, based
				on chief rays. The optional parameter AVG integrates
				over the aperture. Since many rays may be involved (de-
				pending on NRD) in evaluating an average transmission,
				the computing time may increase considerably. If neces-
				sary, reduce NRD to reduce computing time.

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	Weighting Factors for Standard Cameras							
$\lambda(nm)$	$W_{blue}(\lambda)$	$\lambda(nm)$	$W_{green}(\lambda)$	$\lambda(nm)$	$W_{red}(\lambda)$			
370.00	1.00	470.00	1.00	550.00	1.00			
380.00	1.00	480.00	1.00	560.00	1.00			
390.00	3.00	490.00	1.00	570.00	1.00			
400.00	7.00	500.00	2.00	580.00	2.00			
410.00	10.00	510.00	4.00	590.00	3.00			
420.00	12.00	520.00	5.00	600.00	4.00			
430.00	12.00	530.00	8.00	610.00	6.00			
440.00	13.00	540.00	15.00	620.00	8.00			
450.00	13.00	550.00	25.00	630.00	12.00			
460.00	12.00	560.00	13.00	640.00	19.00			
470.00	8.00	570.00	13.00	650.00	22.00			
480.00	4.00	580.00	9.00	660.00	16.00			
490.00	2.00	590.00	2.00	670.00	4.00			
500.00	1.00	600.00	1.00	680.00	1.00			
510.00	1.00							

Table 17.1: Weighting factors for colour contribution index calculation of standard cameras

# **Polarization Analysis**

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Polarization analysis in OpTaliX uses an extension to the classical ray trace, such that vector properties are associated to rays. Interaction at surfaces in the optical system alter these vector properties, like the polarization state.

	Activates/deactivates polarization ray trace
POL YESTIO	yes : enables polarization ray trace for all subsequent analysis
POL YIN	no : disables polarization ray trace
POL LAM	Polarization analysis vs. wavelength.
POL APE	Calculates the degree of polarization for all rays across the pupil.
POL ELL	Plots polarization ellipses for all rays across the pupil.
POR	Polarization raytrace with user-defined rays (e.g. those rays which
	have been previously defined by the SET RAY or SET FAN com-
	mands. )
PA1 x1 y1 phase1	Polarization amplitude and phase components of electric vector 1.
	The phase is given in radians.
PA2 x2 y2 phase2	Polarization amplitude and phase components of electric vector 2.
	The phase is given in radians. This vector is required to define un-
	polarized or partially polarized light. For strictly monochromatic (co-
	herent) radiation, PA2 will not be used in polarization calculations.
	Polarization state of input radiation:
POLSTATE 0 1	0 = unpolarized, uses both vectors PA1 and PA2,
	1 = completely polarized, uses vector PA1 only.
POLRAY [fij	Polarization ray trace. See detailed description in sect. 18.1
wij sij	
zij]	

# **18.1** Tracing a Polarization Ray

Polarization ray tracing is similar to tracing a single ray as given by the RSI and SIN commands (see page 240 for reference).

The commands POLRAY respectively PRSI trace a single ray through the optical system and output the polarization state (X/Y-amplitudes, phase, degree of polarization) associated with this ray. The input polarization is defined by the PA1 and PA2 commands (see also sect. 18.2).

The command syntax is:

prsi [ si..j | gk | wi..j | zi..j | fi..j ] ape\_relX ape\_relY

where ape\_relX and ape\_relY are the relative coordinates of the ray in the entrance pupil. Example:

pa1 0 1 0	! Linear input polarization, oriented along Y-axis
polstate 1	! Assume coherent (completely polarized) radiation
prsi fl si O O	! Trace polarization ray at field f1, image surface si, for chief ray
	(relative pupil apertures 0/0)

A typical output in the text window is:

```
SINGLE RAY POLARIZATION COMPONENTS :
   _____
Field = 1 OBX =
Colour = 1 WL =
                     0.00000 OBY = 546.000 nm
                                           0.00000
 # Pol.Degree
                                  Phasel
                 X1
                            Y1
 1
     1.00000
                0.000000 1.000000
                                    0.0
      1.00000
                0.684547 0.728969
 2
                                      86.4
 3
      1.00000 0.684547 0.728969
                                    86.4
```

# **18.2 Defining Input Polarization**

In order to perform polarization calculations, the polarization properties of the input beam must be fully specified. Any polarization state of input radiation may be expressed by two independent linearly polarized waves with their electric vectors vibrating in two mutually perpendicular directions at right angles to the direction of propagation. Fig. 18.1 shows the polarization vectors associated to a ray.



Figure 18.1: Definition of polarization vectors, a) mutually perpendicular electric vectors, b) polarization vectors attached to a ray.

It is preferable to align the electric vectors  $a_1$ ,  $a_2$  along the (x,y) coordinate axes of an arbitrarily chosen coordinate system, typically the one which is used to describe the optical system. The polarization vectors are then  $a_1 = (0, 1)$  and  $a_2 = (1, 0)$ . For coherent, i.e. strictly monochromatic radiation (POLSTATE 1), the polarization state is always 100% and one vector  $(a_1)$  is sufficient.  $a_2$ will be ignored for this case.

The state of polarization is best represented by the coherency matrix J of the light wave as found for example in Born and Wolf [4]. The coherency matrix is defined as

$$\mathbf{J} = \begin{bmatrix} \langle a_1^2 \rangle & \langle a_1 a_2 e^{i(\Phi_1 - \Phi_2)} \rangle \\ \langle a_1 a_2 e^{-i(\Phi_1 - \Phi_2)} \rangle & \langle a_2^2 \rangle \end{bmatrix} = \begin{bmatrix} J_{xx} & J_{xy} \\ J_{yx} & J_{yy} \end{bmatrix}$$
(18.1)

where  $\Phi$  is the phase difference between the components of each vector. The diagonal elements of **J** are real and are seen to represent the intensities of the components in the x- and y-directions. The non-diagonal elements are in general complex, but they are conjugates of each other. The form of the coherence matrix **J** can be expressed in a simple manner for some cases of particular interest:

#### **18.2.1** Completely unpolarized (natural) light:

Light which is most frequently encountered in nature has the property that the intensity of its components in any direction perpendicular to the direction of propagation is the same. The coherence matrix of natural light of intensity  $I_0$  is

$$\frac{1}{2}I_0 \left[\begin{array}{cc} 1 & 0\\ 0 & 1 \end{array}\right] \tag{18.2}$$

#### **18.2.2** Completely polarized light:

If we suppose that the light is strictly monochromatic, the amplitudes  $a_1$  and  $a_2$  and the phase factors  $\Phi_1$  and  $\Phi_2$  do not depend on the time. In particular, the matrices

$I\left[\begin{array}{rrr}1&0\\0&0\end{array}\right],$	$I\left[\begin{array}{cc} 0 & 0 \\ 0 & 1 \end{array}\right]$
--------------------------------------------------------	--------------------------------------------------------------

each represent linearly polarized light of intensity I, with the electric vector in the x-direction  $(a_2=0)$  and the y-direction  $(a_1=0)$  respectively. For circularly polarized light the coherency matrix is

$$\frac{1}{2}I\left[\begin{array}{cc}1&\pm i\\ \mp i&1\end{array}\right]$$

where I is the intensity of the light. The upper and lower sign is taken according whether the polarization is right- or left-handed.

#### **18.2.3** Some equivalent representations:

We note some useful representations of *natural light*. The coherency matrix of natural light may always be expressed in the form

$$\frac{1}{2}I\begin{bmatrix}1&0\\0&1\end{bmatrix} = \frac{1}{2}I\begin{bmatrix}1&0\\0&0\end{bmatrix} + \frac{1}{2}I\begin{bmatrix}0&0\\0&1\end{bmatrix}$$
(18.3)

and this implies that a wave of natural light, of intensity I, is equivalent to two independent linearly polarized waves, each of intensity  $\frac{1}{2}I$ , with their electric vectors vibrating in two mutually perpendicular directions at right angles to the direction of propagation.

Another useful representation of natural light is

$$\frac{1}{2}I\begin{bmatrix}1&0\\0&1\end{bmatrix} = \frac{1}{4}I\begin{bmatrix}1&+i\\-i&1\end{bmatrix} + \frac{1}{4}I\begin{bmatrix}1&-i\\+i&1\end{bmatrix}$$
(18.4)

and implies that a wave of natural light of intensity I is equivalent to two independent circularly polarized waves, one right-handed, the other left-handed, each of intensity  $\frac{1}{2}I$ .

Thus, for the determination of the polarization behaviour of an optical system, **two** linearly polarized waves (represented by rays) according eq. 18.3 are traced independently through the optical system. The vibrating planes of this incident waves (represented by rays) can be defined by proper setting of the amplitudes  $a_1, a_2$  and the phase difference  $\delta$  between the components  $a_1, a_2$  of each wave.

# **18.3** The Degree of Polarization:

The ratio of the intensity of the polarized portion of the total light intensity is called the *degree of polarization*  $\mathbf{P}$  of the wave. Calculation of  $\mathbf{P}$  requires two mutually perpendicular electric vectors as shown in Fig. 18.1. Two forms of expressing (calculating)  $\mathbf{P}$  are shown below.

#### **18.3.1** Polarzation expressed by Coherence Matrix

On the basis of the *coherence matrix* the degree of polarization is given by

$$\mathbf{P} = \frac{I_{pol}}{I_{tot}} = \sqrt{1 - \frac{4|\mathbf{J}|}{(J_{xx} + J_{yy})^2}}$$
(18.5)

where  $|\mathbf{J}|$  is the determinant of the coherence matrix as given in eq. 18.1 :

$$|\mathbf{J}| = J_{xx}J_{yy} - J_{xy}J_{yx} \ge 0 \tag{18.6}$$

#### 18.3.2 Polarization expressed by Stokes Vectors

The degree of polarization may also be expressed using Stokes vectors

$$P = \frac{\sqrt{s_1^2 + s_2^2 + s_3^2}}{s_0} \tag{18.7}$$

where the Stokes vector is defined by:

$$s_{0} = \langle a_{1}^{2} \rangle + \langle a_{2}^{2} \rangle$$

$$s_{1} = \langle a_{1}^{2} \rangle - \langle a_{2}^{2} \rangle$$

$$s_{2} = 2 \langle a_{1}a_{2}cos\delta \rangle$$

$$s_{3} = 2 \langle a_{1}a_{2}sin\delta \rangle$$
(18.8)

# **18.4** Total Internal Reflection

The *Fresnel formulae* do not apply for total internal reflection. This is the case when light is propagated from an optically denser medium into one which is optically less dense and when the law of refraction

$$\sin\theta_t = \frac{\sin\theta_i}{n_{12}}n_{12} = \frac{n_1}{n_2}$$

does not give a real value for the angle of refraction  $\theta_t$ . The intensity of light which is totally reflected for each component (TE- or TM-wave) is equal to the intensity of the incident light. But the two components are seen to undergo phase jumps of different amounts.

The changes of the phases  $\delta_s$ ,  $\delta_t$  of the components of the reflected and the incident wave can be expressed as [4]

$$\tan\frac{\delta_s}{2} = -\frac{\sqrt{\sin^2\theta_i - n^2}}{n^2\cos\theta_i} \tag{18.9}$$

$$\tan\frac{\delta_t}{2} = -\frac{\sqrt{\sin^2\theta_i - n^2}}{\cos\theta_i} \tag{18.10}$$

where  $n = n_2/n_1$ . Linearly polarized light will in consequence become elliptically polarized on total reflection. The relative phase difference is  $\delta = \delta_s - \delta_t$ .

# Optimization

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Optimization of an optical system requires the solution of a highly nonlinear problem. It is the process by which the aberrations of a lens are minimized by changing selected lens data (*variables*). A *merit-function* is defined by commands relating to different classes of aberrations (e.g. spot diameter, distortion, etc) and constraints to be fulfilled exactly (e.g. focal length, overall length, etc). In order to optimize a system, both merit-function and variables must be defined. All entries in the merit-function must be computable functions of the variables.

Three types of optimization algorithms are available

- **KT** local optimization, minimizes an error function by a damped-least-square (DLS) method subject to solving constraints using Lagrange multipliers and application of the Kuhn-Tucker optimality condition,
- LM local optimization, minimizes an error function using a modified Levenberg-Marquardt algorithm,
- GO global optimization based on an algorithm proposed by M. Isshiki [67].

A brief overview of the algorithms is given in sections 19.1 to 19.3. For a detailed understanding, the reader is referred to the references cited in the corresponding sections.

In order to set up a local optimization (LM, KT), variables, targets and constraints must be defined. This is performed in several steps:

- VAR : Define variables for non-zoomed and zoomed system. See sect. 19.4 for details.
- TAR : Define target functions and constraints, as described in sect. 19.6.
- OPT: Run the optimization (sect. 19.10).

# **19.1 KT-Optimization**

The KT-optimization minimizes an error function by a damped-least-square (DLS) method subject to exactly solving constraints using Lagrange multipliers. The *Kuhn-Tucker*<sup>1</sup> optimality criteria are applied at each iteration to secure that the true local minimum is found within the domain of constraints given. The Kuhn-Tucker conditions are an extension to the classical DLS method. For further

<sup>&</sup>lt;sup>1</sup>also known as Karush-Kuhn-Tucker condition

reading see Spencer [51] and Feder [11]. Closely following Spencer's treatment, the problem is stated as minimizing

$$\sum_{m=1}^{M} w_m^2 \left( \sum_{j=1}^{J} a_{mj} q_j - d_m \right)^2$$
(19.1)

while at the same time solving the set of linear equations

$$\sum_{j=1}^{J} b_{nj} q_j = e_n, \text{ for } i = 1, \dots, N$$
(19.2)

with

$a_{mj} = \partial g_m / \partial p_j$	derivative on functions to be minimized,
$b_{mj} = \partial h_n / \partial p_j$	derivative on functions to be exactly solved,
$q_j$	= parameter increment,
$d_m$	= function aberration (minimize),
$e_m$	= constraint aberration (solve exactly),
$w_m$	= weight factors,

A solution to this problem, written in matrix form, is given by

$$\left(\mathcal{M}^{T}\mathcal{M} + \mathcal{CI}\right)q - \mathcal{B}^{T}\lambda = \mathcal{M}^{T}r$$
(19.3)

with

$\mathcal{M} = \mathcal{W} \mathcal{A}$	= weighted derivative matrix (minimize)
p	la significa austria (a las areatla)
В	= derivative matrix (solve exactly)
${\mathcal I}$	= identity matrix
$\mathcal{C}$	= dumping factor
$r = \mathcal{W}d$	= weighted aberration
$\lambda$	= Lagrange multipliers

At each iteration, that is after solving the set of DLS equations as given in eq. 19.3, the  $1^{st}$  order (necessary) Kuhn-Tucker conditions, which satisfy the optimum solution of a non-linear problem subject to constraints, are then checked:

$$I \qquad \frac{\partial L}{\partial p_j} = \frac{\partial g}{\partial p_j} - \lambda \frac{\partial h}{\partial p_j} = 0 \quad \text{stationary point}$$

$$II \qquad h(p) \le 0 \qquad \qquad \text{feasibility} \qquad (19.4)$$

$$III \quad \lambda h(p) = 0 \qquad \qquad \text{complementary slackness}$$

$$IV \quad \lambda > 0$$

# **19.2 LM-Optimization**

The problem is solved subject to bounds on the variables using a modified Levenberg-Marquardt algorithm and a finite difference Jacobian [10, 30, 35]. The problem is stated as follows:

$$min_{x \in \mathbb{R}^n} \frac{1}{2} F(x)^T F(x) = \frac{1}{2} \sum_{i=1}^m f_i(x)^2$$
(19.5)

where  $m \ge n$  and  $f_i(x)$  is the i-th component function of F(x). From a current point, the algorithm uses the trust region approach and a new point  $x_n$  is computed as

$$x_n = x_c - \left[J(x_c)^T J(x_c) + \mu_c I\right]^{-1} J(x_c)^T F(x_c)$$
(19.6)

 $F(x_c)$  and  $J(x_c)$  are the function values and the Jacobian evaluated at the current point  $x_c$ , respectively. This procedure is repeated until the stopping criteria are satisfied.

#### **19.3** Global Optimization (GO)

The LM- and KT-optimizations presented in the previous chapters are based on damped-least-squares (DLS) methods which, a priori, only finds local minima close to the starting point. The DLS algorithm is not able to find out of a local minimum to obtain other solutions because the damping factor forces the design within that minimum.

Masaki Isshiki [67] proposed a method to escape from a local minimum in order to find other solutions. This function is defined as

$$f_E = \sqrt{H} \cdot exp\left[ -\frac{1}{2W^2} \sum_{j} \mu_j^2 \cdot (x_j - x_{jL})^2 \right]$$
(19.7)

where:

 $f_E$  = escape function, an additional error function

H = height of the escape function

W = width of the escape function

 $x_i$  = the j-th design parameter

 $x_{jL}$  = the value of the j-th parameter at the local minimum

 $\mu_j$  = the scale factor for the j-th design parameter



Figure 19.1: Escape function to increase the merit function.

The escape function  $f_E$  is treated as an additional error function to the merit function of the local optimization. It shall increase the value of the local merit function in the vicinity of the local minimum so that possibly the design can "escape" from the local minimum.

The parameters H and W are crucial in effectively modifying the merit function. H raises the merit function at the local minimum and W gives the approximate range in which the escape function is effective. There is a third parameter T, the distance threshold between solutions, that affects the behaviour of the global optimization.

A new solution is found when the distance  $D_E$  between solutions in the parameter space is greater than an appropriate threshold T. This distance between solutions is defined by:

$$D_E = \sqrt{\sum_{j=1}^{n} \mu_j^2 \cdot (x'_j - x_j)^2}$$
(19.8)

where  $x'_j$  and  $x_j$  are the values of the *j*-th parameter of the two solutions. The designer must set an appropriate threshold *T* for the distance. A new solution is only accepted (and filed) if the distance  $D_E$  is greater than *T* to avoid a design which is essentially the same as the previous design. A low value of *T* creates solutions which are similar in shape, while larger values of *T* will create (fewer) solutions that are more independent of each other.

The problem is that the appropriate initial values for H, W and T are not known when starting the global optimization. The following empirical rules may help in setting reasonable start values:

- The initial value of H shall be approximately the size of the error function that was obtained in the local optimization. The program first calculates the merit function from the local optimization and then sets H = meritfkn. This is the start value for H in the global optimization.
- The initial value of W can be safely set to 1.
- A distance threshold in the range 0.1 < T < 10 is advised. Low values of T create more solutions of similar shape, high values of T create fewer, but more independent solutions
- The merit function and its constraints must be well defined so that the local optimization safely converges, i.e. the local optimizer must not diverge, must not lead to infeasible solutions or violate optical laws. It is advisable that you first locally optimize your optical system. The parameters and constraints of your merit function will then also used in the global optimization.

Entering and defining the global optimization parameters H, W and T is described in sect. 19.15.2. A worked example of a global optimization is given in sect. 19.16.

# **19.4 Editing Variables**

Construction parameters that shall be variable in the optimization can be defined and edited in various ways, in

- the command line
- the surface editor
- in a special spreadsheet like dialog box.

#### **19.4.1** Editing Variables in the Command Line

In the command line, optimization variables may be added or deleted by the commands:

EDI VAR	The EDI VAR command (without parameters) invokes a dia- log box for editing optimization variables (zoomed and non- zoomed) and targets/constraints. See also sect. 19.4.3 for a detailed description of this dialog box. It contains the most commonly used types of optimization variables, however, vari- ables not found in this dialog box must be set or deleted from the command line (see commands below)
VAR sij sk vstr1 vstr2 VARZ sij sk vstr1 vstr2	Add one or multiple variable(s) on surface(s) sij sk de- scribed by vstr1, vstr2, etc. The VAR command is used for single position (non-zoomed) variables, the VARZ form is used for zoomed variables. Multiple variables on a surface may be com- bined in a single line.Examples: var s4 cuy! curvature (CUY) on surface 4 is variablevar s34 cuy thi! curvature and thickness on sur- faces 3-4 are variable.
DEL VAR sij sk vstr1 vstr2	Delete a fixed (non-zoomed) variable described in vstr1, vstr2, etc on surface(s) sij. Example: del var s3 thi! deletes thickness variable on surface 3.
DEL VARZ sij sk vstr1 vstr2 DEL VAR ALL	Delete a zoom variable described in vstr1, vstr2, etc on surface(s) sij. Example: del varz s3 thi ! deletes (zoomed) thickness variable on surface 3. Delete all fixed (non zoomed) variables on all surfaces in the
DEL VARZ ALL	System.         Delete all zoomed variables on all surfaces in the system.

From the main menu, *Optimization / Variables, Constraints*, edit variables/constraints in a spreadsheetlike dialog box. Optionally use the command EDI VAR or click on the VAR tool button in the main window to open the variables/targets dialog.

# 19.4.2 Editing Variables in the Surface Editor

A user friendly way to define and edit optimization variables is done in the surface editor. There is an empty field right to each parameter value which can be used to make it variable in the optimization. Fig. 19.2 shows an example. To make a parameter variable, enter a "v"-character (without the quotes) into the field, for a zoomed parameter a "z" character must be used.

# **19.4.3** Editing Variables in a Dialog Box

A third way to define and edit optimization variables and constraints is via the spreadsheet-like dialog. It is invoked by the EDI VAR command (without any further parameters). A typical layout of the variables/constraints spreadsheet isgiven in Fig. 19.3.

The titles of the variables columns are consistent with the variables descriptions in the table given in Fig. 19.3. Thus, checking a surface in the CUY column makes the curvature of this surface variable. THI is a variable thickness (axial separation), K denotes a variable conic constant, etc.

🌾 Surface Editor: 0:\optalix\examples\Optimization\Zoom-Lens_0.0TX												
Standard Data Decenter, Tilts Asphere GRIN Solves Special Apertures Hologram Misc. Array												
	TYPE	Radius		Distance		GLASS		APE-Y	×.	Shape	GIb	T ^
4	S	66.7030000	$\langle \rangle$	4.254000		LAFN21		26.284	0	circular	0	
5	S	160.779000	۷	1.330000	z			26.024	0	circular	0	
6	S	173.988000	۷	1.400000		LAK9		11.843	0	circular	0	
7	S	16.6530000	V	4.664000		$\mathbf{N}$		9.908	0	circular	0	
				\ ~		zoomed var	iab	le				

fixed variables

Figure 19.2: Editing optimization variables in the surface editor. The curvatures at surfaces 4-7 are (fixed) variables, indicated by "v", the distance of surface 5 is a zoomed variable, marked by "z"

# **19.5** Definition of Variables (VAR)

Variables are defined and edited by the command "EDI VAR". This command applies for both zoomed and non-zoomed variables. A dialog box will be opened.

In case of a multi-configuration (zoom) system,  $\mathbf{n}$  variables will be created internally for each zoomed variable, if n is the number of positions.

Basically, any lens parameter, which can be changed on the command line, may be used as a variable in the optimization. A concise (but not complete) list of variables is given in the following table.

CUY	curvature
CUX	curvature X (toric deformation)
THI	thickness
THR	reference thickness
DEF	defocus
K	conic constant
А	aspheric parameter, $h^4$ for even asphere, $h^2$ for odd asphere
В	aspheric parameter, $h^6$ for even asphere, $h^3$ for odd asphere
С	aspheric parameter, $h^8$ for even asphere, $h^4$ for odd asphere
D	aspheric parameter, $h^{10}$ for even asphere, $h^5$ for odd asphere
Е	aspheric parameter, $h^{12}$ for even asphere, $h^6$ for odd asphere
F	aspheric parameter, $h^{14}$ for even asphere, $h^7$ for odd asphere
G	aspheric parameter, $h^{16}$ for even asphere, $h^8$ for odd asphere
Н	aspheric parameter, $h^{18}$ for even asphere, $h^9$ for odd asphere
ADE	tilt around X-axis
BDE	tilt around Y-axis
CDE	tilt around Z-axis
XDE	X-decenter
YDE	Y-decenter
ZDE	Z-decenter
GZO	gradient Z-offset
DVO	Dispersion offset
DNO	Index offset
GLA	Combined variable, simultaneously makes DNO and DVO variable
	continued on next page

continued from previous page		
Н2	Hologram coefficient 2 (h-term for symmetric HOE, linear x-term for asym-	
	metric HOE)	
HЗ	Hologram coefficient 3 ( $h^2$ -term for symmetric HOE, linear y-term for asym-	
	metric HOE)	
Н4	Hologram coefficient 4 ( $h^3$ -term for symmetric HOE, $x^2$ -term for asymmetric	
	HOE)	
Н5	Hologram coefficient 5 ( $h^4$ -term for symmetric HOE, $x \cdot y$ -term for asymmetric	
	HOE)	
H6	Hologram coefficient 6 ( $h^5$ -term for symmetric HOE, $y^2$ -term for asymmetric	
	HOE)	
Н7	Hologram coefficient 7 ( $h^6$ -term for symmetric HOE, $x^3$ -term for asymmetric	
	HOE)	
Н8	Hologram coefficient 8 ( $h^7$ -term for symmetric HOE, $x^2 \cdot y$ -term for asymmetric	
	HOE)	
Н9	Hologram coefficient 9 ( $h^8$ -term for symmetric HOE, $x \cdot y^2$ -term for asymmetric	
	HOE)	
H10 to H28	Hologram coefficients 10 to 28	
HX1	x-coordinate of object point source for 2-point HOE	
HY1	y-coordinate of object point source for 2-point HOE	
HZ1	z-coordinate of object point source for 2-point HOE	
HX2	x-coordinate of reference point source for 2-point HOE	
HY2	y-coordinate of reference point source for 2-point HOE	
HZ2	z-coordinate of reference point source for 2-point HOE	
Uxx	Coefficients of user-defined surfaces, SPS-ODD surfaces and SPS-XYP sur-	
	faces. 'xx' denotes the corresponding coefficient number. Example: VAR s4	
	U7	
Zxx	Coefficients of Zernike surfaces. 'xx' denotes the corresponding coefficient	
	number. Example: VAR s4 Z7	

# **19.6** Targets and Constraints (TAR)

Optimization requires a set of targets and constraints which are minimized or solved. Targets are, for example, a minimum spot diameter (SPD) or minimum lateral chromatic aberration (LAC). A constraint is a parameter, which is held exactly or shall be greater or smaller than a specified value. For example, holding the focal length (EFL) to a precise value is a constraint.

The entity of the targets and constraints builds up the "merit-function". There is no built-in default merit function. To define a merit function almost any OpTaliX command may be used. Entries to the merit function may be quite complex as arithmetic expressions (such as 2\*sqrt(2)/3), variables (such as \$x) and lens database items (thickness, radius of curvature, etc.) may also be used for defining targets. The commands can be linked with operands and target values. Allowable operands are:

- = Constrains exactly to target value.
- > The target value of the constraint is defined as a minimum value, or lower boundary.
- < The target value of the constraint is defined as a maximum value, or upper boundary.

Target values to be minimized do not require an operand. A short example illustrates typical merit function definitions:

🖗 Variables / Targets	
Common         Zoom           CUY         THI         THR         K         K.x         A         B         C         D         E           OBJ         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I         I	Targets / Constraints Select a target function from the menu or enter targets/constraints directly into the editor field. ▼ Add ef1 = 25 cy s8 f2 w1 0 0 = 0 spd 0
Delete all Variables Glass boundaries Opt Parameters CAM Parameters	Optimize Help Apply Close Run CAM

Figure 19.3: Editing optimization variables in a spreadsheet like dialog box, invoked by the command EDI VAR.

EFL = 100.	The focal length (EFL) shall be exactly 100 mm.
SPD 0	Minimizes spot diameter with target value 0. Since no field, wavelength or zoom parameters are specified, the spots are minimized for <i>all</i> wavelengths, fields and zoom positions.
SPD f23 w4 0	As above, minimizes spot diameter with target value 0. However, spots are minimized only for fields 2 to 3 and wavelength number 4.
! This is a comment line	Comments are indicated by the exclamation mark "!". The rest of the line is then ignored. In blank lines, the excla- mation mark must be the first character of the line. This way, it is also possible to enable or disable selected target functions.
WAV f1 0 ! wavefront	Minimizes rms-wavefront at field 1. The comment right to the exclamation mark is ignored.
SPD F3 Z2 0 ; wt = 0.7	Minimizes spot diameter for field no.3 and zoom position 2. The target value is 0, the relative weight is 0.7.
SPD F4 0	Minimizes spot diameter for field no.4 and all wavelengths. Because no weight is specified, the default weight 1.0 is assumed.

From the list of target definitions, the merit function is then constituted by the weighted sum of "aberrations", i.e. the difference of actual value of the correction status and its specified target value. The actual value of the merit function can be printed by the ERRF command (see page 372). Generally, a more detailed merit function will be required to fulfill specific needs.

The targets/constraints can be defined on the command line directly or in a spreadsheet like dialog.

TAR constraint_condition	Adds a constraint/target to the merit function definition.
	"constraint_condition" is any target/constraint definition
	(see the command examples below).
TAR efl = $100$	Examples of adding a constraint/target to the merit function
TAP $I_{ofl} = 100I$	list. The optimization target, for example "efl = 100",
TAR EII - 100	is given right to the TAR command and may be also en-
TAR spd f1 0	closed in apostrophes.
DEL TAR	Delete all target/constraints definitions in the merit func-
	tion list.

#### 19.6.1 Defining Targets/Constraints in the Command Line

#### 19.6.2 Dialog based editing of Targets/Constraints

The targets and constraints can be defined in a spreadsheet like dialog box, which is invoked from the command line by the command TAR or click on the VAR tool button in the main window. This dialog box is identical to the dialog for variables setting (VAR command), since this dialog offers both settings for variables **and** for targets/constraints.





# **19.6.3** Include Targets from File

Targets may also be included from external files via the #include option. For example,

```
#include mytargets.txt
```

includes target definitions contained in mytargets.txt as if they were written directly in the targets/constraint editor. A file name without path is searched in the directory where the current system resides. Explicitly specify the path if the file to be included shall be searched in a different directory. Any extension is allowed to the file name. #include statements may appear at any place in the targets list, thus, mixed forms of target/constraints expressions and include file declaration are permitted. For example,

```
efl = 100
#include mytargets.txt
spd f1..3 0
```

There is no limit on the number of #include statements, however, nesting of #include is NOT permitted. That is, a file containing target/constraint definitions may not contain #include statements itself.

#### **19.6.4** Targets using Lens Database Items

Targets may also be composed from *lens database items* (see sect. 27), which gives even greater flexibility. A few examples shall illustrate use of lens database items in defining targets/constraints:

thi si-1 = [thi s5]	Requires thicknesses si-1 (the distance before the image
	surface) and thickness 5 to be equal. If thi s5 is a vari-
	able, thi si-1 will be dynamically adjusted as the opti-
	mization process evolves.
thi s7 = [thi s56]	The thickness on surface 7 shall be equal the sum of thick-
	nesses of surfaces 5 to 6.
cy s5 f1 w1 0 1 >	Mix arithmetic instructions with lens database items to
-1/(2*[fno])	build complex targets.

It is advisable to check correctness of target constructions in the command line. For example, the target of the last example in the table above would be queried in the command line (using the EVAluate command, see sect. 26.9, page 464) as

eva -1/(2\*[fno])

When no errors are issued in the text window, the target can be added to the optimization constraints. This example also illustrates that there is no functional difference in command syntax and constraints definition.

In this context it is important to note that square brackets [], which indicate a *lens database item*, are only allowed on the right side of a constraint (i.e. the target to be evaluated). Basically, a lens database item is a function which returns a value. Thus, a constraint assignment such as [thi s5] >  $3 \times [thi s2]$  would assign a number to the left part (thi s5), which would be a contradiction and therefore is not valid. The correct constraint syntax for this example would be: thi s5 >

3\*[thi s2]

#### Notes:

Targets which invoke paraxial parameter should be used with care, for example EFL, BFL, SAP, ... and all third order aberrations. This applies particularly for zoom systems, where the target values will be computed for all zoom positions, if no other qualifier is present. For example, specifying a target "EFL = 50" in a zoom system with two positions used at two focal lengths (say 50 and 100mm), and omitting any other qualifier would attempt the optimization to solve focal length for *all* positions.<sup>2</sup> In such cases it is mandatory to specify the focal length for each zoom position separately. Thus, two distinct constraints must be specified: "EFL z1 = 50" and "EFL z2 = 100". The same logic applies for groups (surface ranges), e.g. EFL s1..4 z3 = 50.

#### **19.6.5** User-defined Constraints

User-defined variables and user-defined functions may also be specified as part of the constraints list. See sections 26.11, 26.16 for the corresponding syntax. Note that user-defined variables must not be confused with optimization variables (such as curvatures, separations, etc.). User-defined variables are only used for storing calculation results and using them in other arithmetic expressions or constraints.

User-defined variables and functions allows the definition of complex constraints which are not found in the list of the built-in constraints. Variables and functions are dynamically updated as the optimization proceeds. For example,

\$x =	5	! Variable assignment
(axxx	== [efl]+[bfl]-\$x	! Defines a complex function.
(axxx	= 100	! Defines a constraint on the function. Note the single "=" sign.

On the examples given above, it is worth to emphasize the difference in using the "==" and "=" operators in optimization constraints. A function definition must use the "==" operator, however, it does not create an optimization constraint. A function statement using the "=" operator constitutes a constraint, i.e. the numeric result of a previously defined function is used as a parameter in the constraint definition.

Constraints on functions accept (<,=,>) operators.

#### 19.6.6 Default Constraints

If enabled, default constraints will automatically be added to the list of target (error) functions. Default constraints are useful for maintaining reasonable dimensions of lenses and air spaces during optimization. For example, default constraints ensure that edge thicknesses are always manufacturable (i.e. greater than a certain fraction of the lens diameter) and that lenses do not intersect (i.e. air edge separation is always positive).

Default constraints avoid the necessity to explicitly specify axial thickness constraints and edge thickness constraints in targets (merit) functions. Default constraints can be enabled or disabled via the DEFC command or in a dialog box, accessible from the main menu *Optimization –> Parameters* and then selecting the 'Default Constraints' tab (see Fig. 19.5, page 360).

Initially, default constraints are disabled. If required, default constraints must be enabled by checking the 'Enable default constraints' check box or by entering DEFC Yes in the command line prior to

<sup>&</sup>lt;sup>2</sup>Absence of a zoom qualifier "z" implies **all** zoom positions).
ę	Optimization Parameters					
	General Levenberg-Marquardt (Ll	M) Kuhn-	Tucker (KT)	Default Constraints	Glass Polygon	Global Opt.
	Enable default constraints	C	nly applied in	n KT-Optimization !		
	Maximum center thickness	MXT 🗌	0.50000	fraction of clear dian	1.	
	Minimum center thickness	MNT	0.10000	fraction of clear dian	1.	
	Minimum edge thickness	MNE	0.10000	fraction of clear dian	1.	
	Minimum axial air space	MNA	0.10000	mm		
	Minimum air edge separation	MAE	0.00200	mm		
	Maximum angle of incidence	MXA 🗌	60.00000	deg. (In preparatio	on )	
	Help Apply	Close	]	Optimize	GO Te	erminate OPT

Figure 19.5: Dialog box for editing default constraints.

executing optimization. Note that default constraints currently only apply to the KT-optimization, they are ignored in the LM-optimization.

Default constraints differ from specific user constraints. Whereas a specific constraint must be explicitly defined and only applies to specific surfaces and/or zoom positions, the default constraints apply to all surfaces and all zoom positions. Default constraints cannot be given different values for different surfaces or different zoom positions. All default constraints are always imposed as bounds and never as equality constraints. default constraints are always controlled with the method of Lagrangian multipliers.

Note that default constraints are only applied to **variable** thicknesses/separations. Non-variable thicknesses are not included to the default constraints list. If a thickness/separation constraint is explicitly defined in the targets (error) function list, that constraint overrides the corresponding default constraint on that surface(s).

Default constraints settings are stored with the prescription data and optimization data for the current optical system in use. This allows individual settings of default constraints for each specific design.

DEFC Yes No	
	Enable (Yes) or disable (No) default constraints handling.
MXT max_ele_center_thi	Constrain maximum center thickness of all variable thickness elements, unless overridden by THI or ET constraints on spe- cific surfaces. MXT is given as a fraction of the maximum clear aperture. The default MXT value is 0.5 * maximum clear aperture.
MNT min_ele_center_thi	Constrain minimum center thickness of all variable thickness elements, unless overridden by THI or ET constraints on spe- cific surfaces. The default MNT value is 1/10 minimum clear diameter.
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MNE min_ele_edge_thi	Constrain minimum edge thickness of all variable thickness el- ements, unless overridden by THI or ET constraints on specific surfaces. The default MNE value is 1/10 minimum clear diame- ter.
MNA min_air_center_thi	Constrain minimum center thickness of all variable air spaces with 'negative' shape (thicker at edge than center), unless over- ridden by THI or ET constraints on specific surfaces. The de- fault MNA value is 0.1mm.
MAE min_air_edge_thi	Constrain minimum edge thickness of all variable air spaces with 'positive' shape (thinner at edge than center), unless over- ridden by THI or ET constraints on specific surfaces. The de- fault MAE value is 0.002mm.
MXA max_angle_inc	Constrain maximum angle of incidence (in degrees) for all ac- tive fields. The default MXA value is 60deg. <b>In preparation!</b>

The default constraints relating to element thickness and spacing are shown in Fig. 19.6. Note that default constraints are only active if the appropriate thicknesses are variable. If a thickness or spacing is frozen (not variable), default constraints on this surface are totally disabled, however, general thickness constraint violations can occur.

#### 19.6.7 Weights on Error Functions

All error function components (targets), except ">" or "<" constraints, can be assigned weights to express a relative importance among the various functions. Weights are arbitrary real numbers of positive value. Arithmetic expressions are not allowed in defining weights. If not specified, the default weight is 1. They can be explicitly overwritten by adding a "WT" qualifier to the specific error function component. For example,

spd 0; wt = 2

assigns the (relative) weight 2.0 to the spot diameter (SPD) function. This means that the relative importance of the spot diameter is two times higher than other functions (aberrations). Weight specifications **must** be separated from the error/target function specification by a semicolon ";".

The following examples explain the concept of "weights" and also show other advanced features:

EFL = 100	Constrains the focal length to exactly 100mm
MFL  s4 = 25	Keep module focal length (defined at surface 4) to 25mm.
bfl > 160.	The (paraxial) back focal length shall be greater or equal to
	160mm
et s34 12.0 > 5.	The edge thickness between surfaces 3 and 4 at height 12mm
	shall be greater/equal 5mm. Note, that edge thickness (ET) is
	also available as a solve parameter. Although this constraint
	will work in optimization (provided there is no ET-solve at the
	corresponding surface), it is advisable to use the solve on ET in
	order to reduce computing load.
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spd f1 0 ; wt = 2	Minimizes spot diameter at field 1. The weight is 2
spd f2 0 ; wt = 1	Minimizes spot diameter at field 2. The weight is 1
spd f3 w13 0 ; wt =	Minimizes spot diameter at field 3 for wavelengths 1 to 3
0.5	
disy f3 0.1	Distortion in Y-direction is minimized to 0.1%. Since there is
	no weight given, the default weight is 1
y f1 w1 s5 0 1 = 0	Constrains the Y-coordinate of a marginal ray (relative pupil co-
	ordinates are $x_p = 0, y_p = 1$ ) at field number 1 and wavelength
	number 1 at surface 5 to zero. Note that all parameters are
	obligatory in order to specify one single ray only. For example,
	omission of the field qualifier (f1) would return Y-coordinates
	for all fields, which can hardly be solved.

## 19.6.8 Weighted Constraints

Weights can also be assigned to constraints which are solved exactly (=). The function is then included in the error function (minimized) instead of being exactly solved. This option should be used sparingly.

WTC weight_on_constraint	Include constraint in the error function (i.e. minimize) in- stead of solving it exactly. Use only with equality con- straints (=).
--------------------------	-------------------------------------------------------------------------------------------------------------------------------------------

The smallest value that achieves control should be chosen. A low value will allow wider deviations from the target. A higher value will achieve a closer approach to the target but more strongly dominates the solution.

Using WTC is not the best way to optimize. It should only be used when targets are far from the present configuration or the exact solution demands a significant change in the optical design. In such cases it is recommended to switch temporarily to LM-optimization. After a sufficiently close point to the targets has been reached, constraints can be exactly solved using the KT-optimization. See also the notes on selecting the best optimization algorithm on page 373.

#### Examples on using weighted constraints (WTC):

efl = 100 ; wtc = 2 efl 100 ; wt = 2

Both forms yield identical results. Note the second form (EFL 100) without the 'equal' qualifier (=). Since it is omitted, the function will be minimized (with relative weight 2) instead of being exactly solved.



#### MNA (minimum axial air space)

Figure 19.6: Default constraints on element thickness and spacings.

# **19.7** Targets/Constraints Overview

EFL [sij   wij   zij]	Equivalent focal length
BFL [ wi   zi ]	Back focal length at used conjugate, wavelength number wi, zoom position zi
SYL [ zi ]	System length (from first surface to last surface, excluding im- age surface)
MAG [zi]	magnification
SAP [zi]	Location of exit pupil from last surface
THI sij	Axial thickness (separation) at surfaces i to j. Example: thi s35 < 5.0
IMD [zk]	Image distance (THI si-1) at zoom position zk. If zk is omit- ted, IMD is calculated at the first zoom position.
	continued on next page

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IMC [zk]	Image clearance, the smaller distance (edge or axis) between surface $i-1$ and the image surface $i$ . Only calculated at zoom position zk. If zk is omitted, the first zoom position is used.
RDY sij	Radius of curvature at surfaces i to j. Example: rdy s5 > 100
OAL [sij]	Overall length, which is the sum of the axial thick- nesses/separations of surfaces i to j. In absence of a surface range specifier, OAL counts from the first surface to the image surface (not to be confused with SYL, which counts from the first surface to the last surface, excluding image surface). Ex- ample: oal $s26 = 50$
AOI sk fi zi wi rel_apeX rel_apeY	Angle of incidence of a ray at surface si, field fi, zoom po- sition zi, wavelength wi. The values rel_apeX, rel_apeY are the relative coordinates in the entrance pupil. The result is in degree. Note that all parameters are obligatory. Example: aoi s3 f5 w1 0 1.
AOR sk fi zi wi rel_apeX rel_apeY	Angle of refraction (or reflection) of a ray with respect to the local surface normal. All parameters, surface sk, field fi, zoom position zi, wavelength wi are obligatory. The values rel_apeX, rel_apeY are the relative coordinates in the entrance pupil. The result is in degree. Example: aor s3 f5 w1 0 1 < 15.
AOE sk fi zi wi rel_apeX rel_apeY	Angle of exit of a ray with respect to the local surface nor- mal. Note that this command is synonymous the the AOR command given above.All parameters, surface sk, field fi, zoom position zi, wavelength wi are obligatory. The values rel_apeX, rel_apeY are the relative coordinates in the en- trance pupil. The result is in degree. Example: aoe s3 f5 w1 0 1 < 15.
X si fi zi wi rel_apeX rel_apeY	Ray X-coordinate at surface si, field fi, zoom position zi, wavelength wi. The values rel_apeX, rel_apeY are the rel- ative coordinates in the entrance pupil. Note that all parameters are obligatory. Example: x s3 f5 w1 0 1 = 10.
Y si fi zi wi rel_apeX rel_apeY	Ray Y-coordinate at surface si, field fi, zoom position zi, wavelength wi. The values rel_apeX, rel_apeY are the rel- ative coordinates in the entrance pupil. Note that all parameters are obligatory. Example: y s3 f5 w1 0 1 = 10
Z si fi zi / wi rel_apeX rel_apeY	Ray Z-coordinate at surface si, field fi, zoom position zi, wavelength wi. The values rel_apeX, rel_apeY are the rel- ative coordinates in the entrance pupil. Note that all parameters are obligatory. Example: z s3 f5 w1 0 1 = 10
CX si fi zi wi rel_apeX rel_apeY	Ray X-direction cosine at surface si, field fi, zoom position zi, wavelength wi. The values rel_apeX, rel_apeY are the relative coordinates in the entrance pupil. Note that all param- eters are obligatory. Example: cx s3 f5 w1 0 1 = 0.1
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CY si fi zi wi	Ray Y-direction cosine at surface si, field fi, zoom position
rel_apeX rel_apeY	zi, wavelength wi. The values rel_apeX, rel_apeY are the
	relative coordinates in the entrance pupil. Note that all param-
	eters are obligatory. Example: cy s3 f5 w1 0 1 = 0.1
CZ si fi zi wi	Ray Z-direction cosine at surface si, field fi, zoom position
rel_apeX rel_apeY	zi, wavelength wi. The values rel_apeX, rel_apeY are the
± ±	relative coordinates in the entrance pupil. Note that all param-
	eters are obligatory. Example: $cz = s3 = f5 = w1 = 0.1$
CXN si	X-direction cosine of vertex surface normal on surface si Ex-
	ample: $cxn s^3 = 0.1$
CYN si	Y-direction cosine of vertex surface normal on surface si Ex-
	ample: $cyn s^3 = 0.1$
CZN ci	7 direction cosing of vertex surface normal on surface of Ex
CZN SI	2-unection cosine of vertex surface normal of surface S1. Ex-
VCC ci	$\frac{1}{1} \frac{1}{1} \frac{1}$
ADC ST	referred to the global coordinate system. If CLO als yes is
	defined the V apprding to is referred to the vertex apprding to of
	defined, the A-cooldinate is felened to the vertex cooldinate of
VCC ci	Vertex V according to of surface of The seconding to return 1.
ISC SI	vertex 1-coordinate of surface s1. The coordinate returned is
	referred to the global coordinate system. If GLO sk—yes is
	defined, the Y-coordinate is referred to the vertex coordinate of
	surface sk. Example: ysc s3
ZSC SI	Vertex Z-coordinate of surface s1. The coordinate returned is
	referred to the global coordinate system. If GLO sk—yes is
	defined, the Z-coordinate is referred to the vertex coordinate of
	surface sk. Example: zsc s3
XSG si	Vertex X-coordinate of surface s1 referred to the global coor-
	dinate system of the system. Use commands XSC and GLO, if
	reference to another (preceding) surface is required.
YSG si	Vertex Y-coordinate of surface si referred to the global coor-
	dinate system of the system. Use commands YSC and GLO, if
	reference to another (preceding) surface is required.
ZSG si	Vertex Z-coordinate of surface si referred to the global coor-
	dinate system of the system. Use commands ZSC and GLO, if
	reference to another (preceding) surface is required.
PATH sij fi zi wi	Physical path-length along a ray between surfaces sij,
rel_apeX rel_apeY	at field fi, zoom position zi, wavelength wi. The values
	rel_apeX, rel_apeY are the relative coordinates in the en-
	trance pupil.
OPL sij fi zi wi	
rel_apeX rel_apeY	Opucal path-length along a ray between surfaces s1], at
	neid II, zoom position zi, wavelength wi. The values
	rel_apex, rel_apeY are the relative coordinates in the en-
	trance pupil. The optical path length is $n \text{ PATH}$ where $n$ is the
	index of retraction at the specified wavelength.
ET sı.j sk height_X	Edge thickness between surfaces si j at surface coordinates
height_Y	(height_X, height_Y).
	continued on next page

continued from previous page	
SPD [wij fij	Spot diameter (rms).
zij]	
SPX [wij fij	Spot diameter (rms), X-section.
SPY [wij fij	Spot diameter (rms), Y-section.
WAV [wij fij	Wavefront aberration (rms).
SPA [zi]	Third order spherical aberration
COMA [zi]	Third order coma
ASTI [zi]	Third order astigmatism
PETZ [zi]	Third order Petzval Sum
DIST [zi]	Third order distortion
LCA [zi]	Third order longitudinal colour
TCA [zi]	Third order tranversal colour
LAC wij [fij	real ray transversal colour
DISX [zij fij]	Distortion (in %) in X-direction
DISY [zij fij]	Distortion (in %) in Y-direction
FDISX [zij fij]	F-Theta distortion (%) in X-direction
FDISY [zij fij]	F-Theta distortion (%) in Y-direction
MTFA [wij zij	Mean value of sagittal and tangential MTF, values range be-
[ fij]	tween 0 and 1. The MTF is computed at the spatial frequency
	defined by the MFR command. Note, that MTF is usually max-
	Imized, that is the target value is 1.
	MIF tangential, values range between 0 and 1. The MIF is
	mend. Note that MTE is usually maximized that is the target
	value is 1
MTES [wi i zi i	MTE sogittal values range between 0 and 1. The MTE is com-
fi il	puted at the spatial frequency defined by the MFR command
	Note that MTF is usually maximized that is the target value is
	1.
UA [sij zij]	Denovial dimetion angle of the manninglamentum new Nates ITA
UMY [sij zij]	and LIMV are supersumers.
HA [si i zi i]	
HMY [sii zii]	Paraxial height of the marginal aperture ray. Note: HA and HMY
	are synonymous.
	Paraxial direction angle of chief ray. Note: UB and UCY are
UCY [S1] Z1]]	synonymous.
HB [sij zij]	Paraxial height of chief ray Note: HB and HCY are synony-
HCY [sij zij]	mous.
WEI [sij]	Weight (in $g/cm^2$ )
MFL	Module focal length
VIG [fk]	Vignetting factor relative to field 1. Values are returned be-
	tween 0 (100% vignetting) and 1 (no vignetting). If fk is omit-
	ted, the maximum field is used.
	continued on next page

continued from previous page	
TSF [fk fij wk wij] sk sij	Tolerance sensitivity on test-plate fit. Note that TSF is the sen- sitivity on DLF tolerance. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLF or a description of test plate fit on page 411. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLF 2.0 (fringes) for calculating tolerance sensitivity TSF.
TSI [fk fij wk wij] sk sij	Tolerance sensitivity on surface irregularity. TSI is the sensitiv- ity on IRR tolerance. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command IRR on page 407. If a tolerance on this parameter has not been defined in the tolerance editor, the program as- sumes IRR 0.4 (fringes) for calculating tolerance sensitivity TSI.
TST [fk fij wk wij] sk sij	Tolerance sensitivity on surface thickness (distance). Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLT on page 407. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLT 0.02 for calculating tolerance sensitivity TST.
TSN [fk fij wk wij] sk sij	Tolerance sensitivity on index of refraction. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining index tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLN 0.001 for calculating tolerance sensitivity TSN.
TSV [fk fij wk wij] sk sij	Tolerance sensitivity on dispersion. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLV $0.008 (0.8\%)$ for calculating tolerance sensitivity TSV.
TSX [fk fij wk wij] sk sij	Tolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLX, page 407, for defining dis- persion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLX 0.02 (mm) for calculating tolerance sensitivity TSX.

continued from previous page	
TSY [fk fij wk wij] sk sij	Tolerance sensitivity on Y-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLY, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLY 0.02 (mm) for calculating tolerance sensitivity TSY.
TSZ [fk fij wk wij] sk sij	Tolerance sensitivity on Z-decenter. A Z-decenter is equiva- lent to a thickness tolerance. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLZ, page 407, for defining dispersion tol- erances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLZ 0.05 (mm) for calculating tolerance sensitivity TSZ.
TSA [fk fij wk wij] sk sij	Tolerance sensitivity on tilt about X-axis. Requires that a tol- erance has been defined on the corresponding surface in the tolerance editor. See the command DLA, page 407, for defin- ing dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLA 5 (arcmin) for calculating tolerance sensitivity TSA.
TSB [fk fij wk wij] sk sij	Tolerance sensitivity on tilt about Y-axis. Requires that a tol- erance has been defined on the corresponding surface in the tolerance editor. See the command DLB, page 407, for defin- ing dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLB 5 (arcmin) for calculating tolerance sensitivity TSB.
TSG [fk fij wk wij] sk sij	Tolerance sensitivity on tilt about Z-axis. Requires that a tol- erance has been defined on the corresponding surface in the tolerance editor. See the command DLG, page 407, for defin- ing dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLG 5 (arcmin) for calculating tolerance sensitivity TSG.
TSH [fk fij wk wij] sk sij	Tolerance sensitivity on index homogeneity. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command HOM, page 407, for defining homogeneity tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes HOM $50 (50 \cdot 10^{-6})$ for calculating tolerance sensitivity TSH.
	continued on next page

continued from previous page	
TSR [fk fij wk wij] sk sij	Tolerance sensitivity on radius change. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLR, page 407, for defining homogeneity tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes a radius change DLR 0.0025 (mm) for calculating tolerance sensitivity TSR.

## 19.8 Controlling Contrast vs. Resolution

Optimizing for spot (SPD) or wavefront (WAV) alone is often not a sufficient criterion for achieving the desired result and a finer adjustment of the spot or wavefront shape may be necessary. In particular, emphasizing the central core of a spot will increase spatial resolution at the expense of a lowered contrast. The WTA command, as described below, allows the designer to balance performance between contrast and resolution.

			Weight on aperture. Controls relative weight given to the center of each ray bundle (high values) vs. the edge. The effect of this parameter is to balance between contrast and resolution. Typical values:				
WTA	[zk]	aperture_weight	weight Conditions				
			0.0 High contrast, good resolution				
			0.5	Good contrast, high resolution			
			1.0	Low contrast, very high resolution.			
			See also exa	imples below.			

The relative weight across the aperture follows the function

$$W = e^{-(WTA \cdot r)^2} \tag{19.9}$$

where r is the relative aperture radius and W is the relative weight (a number between 0 and 1) applied to the ray. This function is similar to the apodization function as described in section 7.3.6 (page 53). The main difference, however, is that WTA is *only* applied to spot or wavefront calculation in optimization, whereas pupil apodization is applied to *all* performance analyses. That is, pupil apodization -if defined- is always in effect, WTA is only used in optimization. Also note that Eq. 19.9 indicates arbitrary WTA values, however, for best performance  $0 \le WTA \le 1$  is recommended.

Figs. 19.7 and 19.8 show the effect of WTA on spot (or wavefront) shape.

## 19.9 Glass Optimization and Glass Map Boundary Points

It is sometimes desirable to let glasses "float" during optimization, i.e. the optimizer selects an appropriate glass in a continuous  $n - \nu$  domain. To accomplish this, the DNO and/or DVO variables at a surface must be activated, which means that index and dispersion may vary during optimization and appropriate n and  $\nu$  offsets are applied to the base glass. Internally, a glass with DNO/DVO offsets is modelled as a fictitious glass. It is, however, necessary to constrain the range in which index n and dispersion  $\nu$  may vary, because otherwise n and  $\nu$  will likely arrive at infeasible points.



Figure 19.7: Effect of 'weight on aperture' (WTA) on spot shape (left) and transverse aberrations (right), by minimizing spot diameter (e.g. spd fl 0). High values emphasize the central core of the spots at the expense of a larger blur.

This range is defined by a **convex** polygon in the standard SCHOTT diagram, describing the outer boundaries of the allowable area in which the glasses must lie. Up to 20 polygon points may be specified. The following diagram shows the default glass polygon which encloses the majority of the SCHOTT glasses:

The error value of a fictitious (floating) glass is defined by the (vertical) distance of the fictitious  $n - \nu$  coordinates from each boundary line. The error values must always be negative in order for the fictitious glass to stay within the glass map boundary polygon.

The glass map boundary ('glass polygon') is specified using the following command syntax:

	Define glass map corner points ("glass polygon"). The glass map bound- ary points can be specified by the following forms:		
GLP corner1	xxx.yyyFictitious glass code. For example 514.643nnnnnnA six-digit glass code. For example 514643predefined glassA 1- to 10-character alphanumeric code from the predefined glass catalogue.		
corner2 n	Mixed forms are permitted. Note that the polygon must be <b>convex</b> and		
or	corners must be specified in clockwise orientation in the $n - \nu$ diagram. Examples :		
GLP DEF	GLP 481.850 820.501 900.234 560.410 481.850 GLP BK7 N-Lak9 SF6 F2 BK7 GLP BK7 683542 SF6 531.422 BK7		
	The alternate form GLP DEF restores the default glass map boundary according to table 19.9.		
EDI GLP	Edit glass map boundaries in a dialog.		

The current setting of the glass map boundaries may be listed by the command LIS GLP. The default glass map boundaries are defined by a 7-point polygon in the  $n - \nu$  domain (see also Fig. 19.9), to



Figure 19.8: Effect of 'weight on aperture' (WTA) setting on MTF. High values improve the high-frequency components of MTF (i.e. high resolution), low values improve the low-frequency components of MTF (i.e. high contrast). Note that the curves above only show the case of improving high-frequency components.

match the domain of current SCHOTT glasses.

#### Notes:

The DNO and DVO variables are understood in a continuous  $n - \nu$  domain, in contrast to the fixed properties of real glasses. Thus, n and  $\nu$  offsets are fictitious additives to the currently selected glass. The dispersion offset is modelled as a fictitious MIL-glass which lies perfectly on the so-called Abbeline ("normal" line).

A glass map polygon must be closed, that is, the last corner must be identical with the first corner.

Fictitious glasses obtained after an optimization run can be converted to a regular catalogue glass by the REG command (see also page 200). This option searches for the nearest catalogue glass on the basis of the DNO/DVO offsets and automatically replaces the continuous glass model by a fixed catalogue model. The REG option, however, does not eliminate DNO/DVO variables on that glasses.

Point	$n_d$	$ u_d$
1	87.00	1.4800
2	41.00	1.8900
3	20.00	1.9300
4	25.00	1.7700
5	37.00	1.5700
6	57.00	1.4900
7	87.00	1.4800

Table 19.9: Default glass map boundaries matched to SCHOTT glasses.



Figure 19.9: Definition of default glass map boundary.

# **19.10** Run the Local Optimization (OPT)

Once variables, targets and constraints are defined, the optical system can be locally optimized.

OPT [LM   KT   n_steps   SIL]	Run the <b>local</b> optimization. The optional parame- ters LM, and/or KT specify the algorithm to be used. $n\_step$ defines the maximum number of optimization steps (iterations) and SIL switches to <b>silent</b> mode, i.e. any output is suppressed. See also the guidelines for se- lecting the appropriate algorithm. If neither LM, nor KT is specified, the selected method of the previous opti- mization run is repeated. Initially, KT-optimization will be used. If no parameter is given, the default number of iterations is p_stops = 10
LINDO OPT	Undo last optimization i.e. it restores the state of the
	optical system before the optimization. This command is particularly useful if the optimization run failed to converge. For example, ill-conditioned or contradictory constraints will often lead to infeasible conditions. Undo is a one-step operation, i.e. only the last optimization can be undone.
ERRF	Print detailed error (merit) function including the error contributions of each constraint. This is a diagnostic tool to identify the most disturbing aberrations. It does not run the optimization.

opt		! initially uses KT-optimization, otherwise the method from the previous ! optimization run is repeated.
opt ln	n 5	! uses LM-optimization, stop after 5 iterations.
opt ln	n kt 10	! LM- and KT-optimization are executed successively, 10 iterations each,
opt kt	-	! KT-optimization only.
opt si	il	! Silent optimization (no output).

#### Examples:

#### 19.10.1 Selecting the appropriate local Optimization Method

As described in sections 19.1, 19.2, OpTaliX provides two different optimization methods (KT- and LM optimization), and the question may arise which method is preferred under certain conditions. This section describes the pros and cons of each method and attempts to give recommendations for various cases.

The **Kuhn-Tucker** (**KT**) algorithm solves constraints (i.e. =, >, < operations) exactly, while other functions are solved in a least-squares sense. It provides precise control of the constraints and it is not necessary to choose appropriate weights for each constraint and modifying it as the design process evolves. However, the user may (temporarily) overrule exact solving of equality constraints by the WTC command, which converts behaviour of the KT-optimization only for that specific constraint similar to properties of the LM-optimization (i.e. weighting that constraint).

If lens parameters are to be exactly controlled, for example object-image distance OAL, the KToptimization gives *exact* solutions. Due to the highly non-linear nature of almost all aberrations in optical systems, it takes a few iterations to accurately control the desired parameters.

In the hands of an inexperienced user, however, the KT-optimization may cause difficulties, depending on the problem definition. For example, if a user inadvertently defines incompatible conditions, the resultant equations become indeterminate and optimization will not proceed. In such cases the program issues a warning message and prints the conflicting constraint(s).

Note that KT-optimization is the preferred (default) method in OpTaliX.

Basically, the **Levenberg-Marquardt** (**LM**) algorithm is an unconstrained damped least-squares algorithm. Constraints (i.e. =, >, < operations) are handled like aberrations, except that higher weights are generated internally for these functions. This approach is preferable when the design is at an early stage of development and the optical performance is far from the design goal. In case of improperly defined or even incompatible constraints, it is unlikely that the LM-optimization will destroy the design. Contrary to the KT-optimization, the program will simply find the best compromise between the incompatible conditions. That is, it will rather 'squeeze' the design smoothly into a different form, which in almost all cases is still computable. Boundary conditions (<, >), for example, are not solved precisely, instead they are held very close to the desired target. One particular advantage is that constraints can be given large or small weight, depending on their importance. On the other hand it requires that constraint weights and target weights must be properly balanced to achieve the desired result.

Note that the optimization routines can only solve problems which have been specified by the user. In particular, they cannot

- Violate the law of optics,
- solve for more constraints than the number of variables you have provided,
- Solve for a constraint when there is no variable for it,

- add or remove elements or dramatically re-arrange the optical system,
- control aberrations that are uncorrectable (for examples astigmatism in doublets, distortion in eyepieces).

## 19.10.2 MTF Optimization

Using the modulation transfer function (MTF) directly as target in optimization often leads to unsatisfactory success, particularly to less experienced designers. One major problem with using MTF optimization is the fact that MTF values may oscillate significantly as a function of construction parameters. To illustrate the problem, consider the change of MTF as a function of defocus, i.e. when the image plane is moved forward and backward along the optical axis. Fig. 19.10 indicates the large MTF variation as the image plane is moved away from the optimum position (axial distance = 0). The success of the optimization will now depend on the initial starting point. Assume we have chosen staring point (1), which is at an axial distance  $z \approx 0.6$ , the side maximum will be found, because a locally optimizing algorithm cannot jump over adjacent minima/maxima.



Figure 19.10: Variation of diffraction MTF for a perfect lens as a function of defocus.

A better starting point would be (2) where the optimization algorithm can find the 'true' MTF maximum without intermediate valleys. It is more realistic to use MTF optimization for systems which are close to the optimum and which can benefit from a final tuning. It is therefore good practise to run optimization using spot diameter (SPD) or wavefront variance (WAV) *prior* to optimizing MTF directly.

# **19.11** Optimizing for Tolerance Sensitivity

In the (iterative) design and optimization process it is often wanted not only to reduce aberrations, but also reducing sensitivity for parameters, such as decenter, tilt, thickness tolerances, etc. The driving force are manufacturing issues where manufacturing tolerances as large as possible are desired.

OpTaliX helps you to simultaneously optimize for image performance and tolerance sensitivity on selected parameters, already in the design stage. Tolerance sensitivity is a measure for the change of performance  $\Delta\Phi$  (aberration, merit function) given a certain perturbation  $\Delta x$  of a construction parameter. Therefore, OpTaliX attempts to minimize the tolerance sensitivity function S

$$S = \sqrt{\sum_{i}^{N} \left(\frac{\Delta\Phi}{\Delta x}\right)^2} \tag{19.10}$$

where *i* is the surface number. The performance change  $\Delta \Phi$  is always calculated on the basis of wavefront aberration (WAV) for each tolerance item. It should be noted that optimizing for **both** performance  $\Phi$  and tolerance sensitivity *S* is a contradictory process. It often seems impossible to reduce tolerance sensitivity without sacrificing performance. Generally, a subtle balance between  $\Phi$  and *S* must be selected. Finding this balance is the responsibility and skill of the optical designer. Further information on this subject is also given by Grey [16], and Isshiki et.al, [23].

## **19.11.1** Tolerance Sensitivity Items

OpTaliX provides several commands to calculate tolerance sensitivity, TSF, TST, TSI, TSN, TSV, TSX, TSY, TSZ, TSA, TSB, TSG, as defined in section 19.7 (page 363). These tolerance sensitivity commands assume that an appropriate tolerance has been assigned in the tolerance editor (page 410). If tolerances on requested parameters are not available, respectively not defined in the tolerance option (sect. 22.5, page 417), the program assumes the following parameter changes (tolerances)  $\Delta x$  for calculating tolerance sensitivity:

Item	Effect	Default tolerance
TSF	Sensitivity on surface fit tolerance (DLF)	$\Delta x = 2$ fringes
TSI	Sensitivity on surface irregularity tolerance (IRR)	$\Delta x = 0.4$ fringes
TST	Sensitivity on axial thickness tolerance (DLT)	$\Delta x = 0.1 \text{ mm}$
TSN	Sensitivity on refractive index tolerance (DLN)	$\Delta x = 0.001$
TSV	Sensitivity on dispersion tolerance (DLV)	$\Delta x = 0.008$
TSR	Sensitivity on radius of curvature tolerance (DLR)	$\Delta x = 0.0025$
TSX	Sensitivity on X-decenter tolerance (DLX)	$\Delta x = 0.02 \text{ mm}$
TSY	Sensitivity on Y-decenter tolerance (DLY)	$\Delta x = 0.02 \text{ mm}$
TSZ	Sensitivity on Z-decenter tolerance (DLZ)	$\Delta x = 0.05 \text{ mm}$
TSA	Sensitivity on $\alpha$ -tilt (about X-axis) (DLA)	$\Delta x = 5 \operatorname{arcmin}$
TSB	Sensitivity on $\beta$ -tilt (about Y-axis) (DLB)	$\Delta x = 5 \operatorname{arcmin}$
TSG	Sensitivity on $\gamma$ -tilt (about Z-axis) (DLG)	$\Delta x = 5 \operatorname{arcmin}$
TSH	Sensitivity on homogeneity tolerance (HOM)	$\Delta x = 50 \cdot 10^{-6}$

Commands for defining Tolerance Sensitivity Items			
TSF [fk fij wk wij] sk sij	Tolerance sensitivity on test-plate fit. Assumes that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLF or a description of test plate fit on page 411. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLF 2.0 (fringes) for calculating tolerance sensitivity TSF.		
	continued on next page		

TSI[fk fij] wk wij] sk sijTolerance sensitivity on surface irregularity. Assumes that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command IRR on page 407. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes IRR 0.4 (fringes) for calculating tolerance sensitivity TSI.TST[fk fij] wk wij] sk sijTolerance sensitivity on surface thickness (distance). Requires that a tolerance on this parameter has not been defined on the corresponding surface in the tolerance editor. See the command DLT on page 407. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLT 0.02 for calculating tolerance sensitivity TST.TSN[fk fij] wk wij] sk sijTolerance sensitivity on index of refraction. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining index tolerances. If a tolerance sensitivity TSN.TSV[fk fij] wk wij] sk sijTolerance sensitivity on dispersion. Requires that a tolerance editor. See the command DLN, page 407, for defining index tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLN 0.001 for calculating tolerance. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLV 0.008 (0.8%) for calculating tolerance ensitivity TSV.TSX[fk fij] wk wij] sk sijTolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, see the command DLX, page 407, for defining dispersion tolerances. If a tolerance on this parameter has	continued from previous page	
TST[fk fij] wk wij] sk sijTolerance sensitivity on surface thickness (distance). Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLT on page 407. If a tolerance con this parameter has not been defined in the tolerance editor, the program assumes DLT 0.02 for calculating tolerance sensitivity TST.TSN[fk fij] wk wij] sk sijTolerance sensitivity on index of refraction. Requires that a toler- ance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining index tolerances. If a tolerance on this parameter has not been defined in the tolerance editor. See the command DLN, page 407, for defining index tolerance sensitivity TSN.TSV[fk fij] wk wij] sk sijTolerance sensitivity on dispersion. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLV 0.008 (0.8%) for calculating tolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLX, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLX, page 407, for defining dispersion toler- ances. If a tolerance ensitivity TSV.TSY[fk fij] wk wij] sk sijTolerance sensitivity on Y-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance edi	TSI [fk fij wk wij] sk sij	Tolerance sensitivity on surface irregularity. Assumes that a tol- erance has been defined on the corresponding surface in the toler- ance editor. See the command IRR on page 407. If a tolerance on this parameter has not been defined in the tolerance editor, the pro- gram assumes IRR 0.4 (fringes) for calculating tolerance sensi- tivity TSI.
TSN [fk fij wk wij] sk sijTolerance sensitivity on index of refraction. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining index tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLN 0.001 for calculating tolerance sensitivity TSN.TSV [fk fij wk wij] sk sijTolerance sensitivity on dispersion. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLV 0.008 (0.8%) for calculating tolerance sensitivity TSV.TSX [fk fij wk wij] sk sijTolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLX, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLV 0.008 (0.8%) for calculating tolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLX, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLX 0.02 (mm) for calculating tolerance sensitivity TSX.TSY [fk fij wk wij] sk sijTolerance sensitivity on Y-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLY, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLX 0.02 (mm) for calculating tolerance sensitivity TSX.	TST [fk fij wk wij] sk sij	Tolerance sensitivity on surface thickness (distance). Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLT on page 407. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLT 0.02 for calculating tolerance sensitivity TST.
TSV [fk fij wk wij] sk sijTolerance sensitivity on dispersion. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLV 0.008 (0.8%) for calculating tolerance sensitivity TSV.TSX [fk fij wk wij] sk sijTolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLX, page 407, for defining dispersion toler- 	TSN [fk fij wk wij] sk sij	Tolerance sensitivity on index of refraction. Requires that a toler- ance has been defined on the corresponding surface in the toler- ance editor. See the command DLN, page 407, for defining index tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLN 0.001 for cal- culating tolerance sensitivity TSN.
TSX [fk fij wk wij] sk sijTolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLX, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLX 0.02 (mm) for calculating tolerance sensitivity TSX.TSY [fk fij wk wij] sk sijTolerance sensitivity on Y-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLY, page 407, for defining dispersion toler- calculating tolerance sensitivity TSX.TSY [fk fij wk wij] sk sijTolerance sensitivity on Y-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLY, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLY 0.02 (mm) for calculating tolerance sensitivity TSY.	TSV [fk fij wk wij] sk sij	Tolerance sensitivity on dispersion. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLV 0.008 (0.8%) for calculating tolerance sensitivity TSV.
TSY [fk fij wk wij] sk sijTolerance sensitivity on Y-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLY, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLY 0.02 (mm) for calculating tolerance sensitivity TSY.	TSX [fk fij wk wij] sk sij	Tolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLX, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLX 0.02 (mm) for calculating tolerance sensitivity TSX.
	TSY [fk fij wk wij] sk sij	Tolerance sensitivity on Y-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLY, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLY 0.02 (mm) for calculating tolerance sensitivity TSY.

OpTaliX

continued from previous page	
TSZ [fk fij wk wij] sk sij	Tolerance sensitivity on Z-decenter. A Z-decenter is equivalent to a thickness tolerance. Requires that a tolerance has been de- fined on the corresponding surface in the tolerance editor. See the command DLZ, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLZ 0.05 (mm) for calculating tol- erance sensitivity TSZ.
TSA [fk fij wk wij] sk sij	Tolerance sensitivity on tilt about X-axis. Requires that a toler- ance has been defined on the corresponding surface in the toler- ance editor. See the command DLA, page 407, for defining dis- persion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLA 5 (ar- cmin) for calculating tolerance sensitivity TSA.
TSB [fk fij wk wij] sk sij	Tolerance sensitivity on tilt about Y-axis. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLB, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLB 5 (arcmin) for calculating tolerance sensitivity TSB.
TSG [fk fij wk wij] sk sij	Tolerance sensitivity on tilt about Z-axis. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLG, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLG 5 (arcmin) for calculating tolerance sensitivity TSG.
TSH [fk fij wk wij] sk sij TSR [fk fij	Tolerance sensitivity on index homogeneity. Requires that a tol- erance has been defined on the corresponding surface in the tol- erance editor. See the command HOM, page 407, for defining homogeneity tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes HOM $50 (50 \cdot 10^{-6})$ for calculating tolerance sensitivity TSH.
wk wij] sk sij	Tolerance sensitivity on radius change. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLR, page 407, for defining homogeneity tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes a radius change DLR 0.0025 (mm) for calculating tolerance sensitivity TSR.

## 19.11.2 Using Tolerance Sensitivity Items in Optimization

If optimizing (minimizing) for tolerance sensitivity, the various tolerance sensitivity items described in the previous section should be understood as *aberrations* added to the targets/constraints (merit function) list. The syntax for defining tolerance sensitivity in optimization is found in sect. 27.1, page

483. Here is a typical example in the optimization targets/constraints list:

Focal length shall be exactly 100mm.
Spot diamotor (rms) shall be zero (minimized) for all fields
wavelengths, zoom positions.
Tolerance sensitivity on surface tilt about X-axis shall be minimized for surfaces 1-5, fields 1-2 and wavelength number 1.
Tolerance sensitivity on surface Y-decenter shall be min- imized for <b>all</b> surfaces, <b>all</b> fields and <b>all</b> wavelengths de- fined in the system configuration.

#### Notes:

- Do not attempt to request a tolerance sensitivity item to become exactly zero, e.g. 'TSA = 0' as this is impossible on elements/surfaces that have optical effect. Instead minimize it by omitting the equal '=' sign in the constraints definition, e.g. 'TSA 0'.
- It is generally advisable to start with low weights on tolerance sensitivity constraints, for example

tsa sa f1 0 ; wt = 0.1

By gradually increasing the corresponding weight, an acceptable compromise between performance and general tolerance sensitivity is quickly found.

## **19.12** Description of Output

A typical output from an optimization run is shown below (load  $\phi a link \phi a link \$ 

KT OPTIM	IZATION:							
Number	of variables		: 13					
Number	of functions		: 2754					
Number	of equality cons	traints	: 1					
Number	of inequality co	nstraints	: 4					
Number	of internal cons	traints	: 4					
OPTIMIZA	TION PARAMETERS :							
Number	of iterations	: m	in = 2	max =	15			
ORGR (	Optimization Ray	Grid) : 1	6					
IMPR (	Fractional Improv	ement) : 0	.01000					
WTA (	Weight on Apertur	e) : 0	.00000					
DEFC (	Default Constrain	ts) : Y	es					
Targets/	Constraints		Targe	et	Function	E	rror	Violation
efl = 60			60.0000	0 4	9.999580	-10.00	0420	* *
spd 0			0.0000	00	0.009321	0.00	9321	
Default	Constraints		Targe	et	Function	E	rror	
MAE S6		>	0.00200	0 0	5.274917	5.27	2917	
MXT S7		<	10.14773	16	2.009000	-8.13	8716	
MNT S7		>	2.0295	43	2.009000	-0.02	0543	*
MNE S7		>	2.0295	43	4.229104	2.19	9560	
Iter	Min.	Equal		Inequal.	Dı	umpingF.	Imj	prov.
0	0.398957	3.16234	4	0.143329	1.000	0000		
1	6.332909	1.71054	7	0.000000	1.000	0000	-14.8	87367

2	1.941585	0.635908	0.000000	0.625000	0E-01 0	.69341
3	0.470827	0.452288	0.00000	0.232236	9E-02 0	.75750
4	0.217870	0.145856	0.00000	0.162825	9E-02 0	.53726
5	0.206532	0.144571	0.00000	0.101766	2E-03 0	.05204
6	0.183684	0.066643	0.00000	0.101766	2E-03 0	.11063
7	0.168225	0.075135	0.00000	0.101766	2E-03 0	.08416
8	0.159436	0.158571	0.00000	0.504566	0E-04 0	.05224
9	0.154823	0.011828	0.00000	0.897190	2E-04 0	.02893
10	0.152053	0.022684	0.00000	0.104838	7E-03 0	.01789
11	0.151615	0.013254	0.00000	0.726001	2E-04 0	.00288
Optimiza	tion stopped.	Improvement is less	than 0.01	000 (1.00%	)	
Targets/	Constraints	Ta	rget Fu	nction	Error	Violation
efl = 60	•	60.00	0000 60.	000176	0.000176	
spd O		0.00	0000 0.	004111	0.004111	
Default	Constraints	Ta	rget Fu	nction	Error	
MAE S6		> 0.00	2000 11.	715292	11.713292	
MXT S7		< 10.14	7716 5.	052111	-5.095605	
MNT S7		> 2.02	9543 5.	052111	3.022568	
MNE S7		> 2.02	9543 7.	034676	5.005132	

In the first section a listing of the number of variables and constraints is shown. Equality and inequality constraints are separately listed. Following this is a list of the user-defined constraints with the target-, function- and error-values of the starting system (i.e. prior to optimization).

The last column indicates violations on constraints (i.e. equal, less than or greater than), shown as a bar of asterisks (\*) in steps of 10%. The maximum bar length is ten asterisks corresponding to 100% deviation.

If requested, default constraints are tabulated. These are constraints created internally by the program for all variable thicknesses in order to maintain reasonable minimum/maximum element, air-space and edge thickness dimensions. The DEFC command enables (Yes) or disables (No) default constraints.

Each iteration step outputs the merit functions on constraints to be minimized ('Min.' column), to be held exactly ('Equal.' column), and the inequality ('Inequal.' column) constraints together with the current dumping factor and a relative improvement compared to the previous iteration step. For example, a relative improvement factor 0.01 corresponds to a 1% improvement with respect to the previous iteration. Note that the improvement factor only applies to the KT (Kuhn-Tucker) optimization; it is ignored in the LM (Levenberg-Marquart) optimization.

Iteration terminates if the improvement factor is below a threshold defined by the IMPR command. The error function components of the refined optical system are listed.

#### **19.12.1** List of Active Constraints

Inequality constraints are dynamically added or released during optimization, depending on whether they are violated by a solution or if they are in an acceptable region. When constraints are released they are allowed to drift into the acceptable region without affecting the solution. When constraints are added, the derivatives of the new constraints are calculated and added to the matrix. This causes additional 'minor' solution cycles to be calculated.

Active constraints are only reported if enabled in the Optimization Parameters dialog (there is currently no command line equivalent). From the main menu, select *Optimization* --> *Optimization Parameters* and in the 'Kuhn-Tucker (KT)' tab check 'Show active constraints for each cycle'. A sample output would be

Active Constraints ( 4)	Value	Target	Cost
thi s3 > 8	7.06120	8.00000	-0.415859E+01

thi	s5 > 8	7.50000	8.00000	0.319846E+00
MNE	S3	0.63518	2.40000	0.227979E+02
MNE	S5	1.65757	2.40000	0.359234E+01

The output includes target/boundary values, the actual value and the relative "cost" of imposing the constraints. The relative cost is the "pressure" that a constraint applies to the solution.

Inactive constraints are not included in the 'active constraints' listing. Only if a constraint becomes active, it shows up in the constraints listing.

## **19.13** Terminating Optimization

Optimization is terminated if

- the maximum number of iterations is reached, or
- the "Terminate OPT" button has been pressed in the lower right corner of the optimization parameter dialog (see Fig. 19.11), or
- the fractional improvement of the merit function is below a certain limit value, or
- the number of ray trace errors (if any) has exceeded a certain limit.

The maximum number of iterations is set in the optimization parameter dialog or by the command MXC. See section 19.15 for further information.

Optimization can also be interrupted if ray trace errors occur and a certain number of ray errors has been exceeded. The limit of allowable ray trace errors is set by the OERR command. See sect. 19.15 for details.

The limit on fractional improvement of the merit function is set by the IMPR command. That is, if the improvement of the merit function is smaller than IMPR, optimization will be terminated.

If the ESC-key is pressed, a dialog box will be invoked asking the user whether to terminate or to continue optimization. Note that it may take a while for the dialog to appear because a running iteration step must first be finished. It is therefore recommended to press the ESC-key only once.

A prematurely terminated optimization leaves the optical system in the state of the last iteration step, that is, before the ESC-key was pressed. This state is most likely not the optimum condition (i.e. minimum aberrations), however there are numerous reasons to interrupt optimization (for example, convergence is low, inappropriate variables/constraint settings, time reasons, etc).

## **19.14** Undo Optimization

Optimization can be "undone" by selecting from the main menu *Optimization -> Undo last optimization step*, or from the command line

UNDO OPT

Note that "undo" only applies to the *last* optimization run. Multiple subsequent optimization cycles (prior to the last cycle) cannot be undone. It is recommended to save promising solutions in separate files.

## **19.15** Optimization Parameters

Dialog based editing of optimization parameters is accomplished from the main menu, *Optimization*  $\rightarrow$  *Parameters*. The dialog box as shown in Fig. 19.11 contains several tabs. In the main (general) tab, the optimization algorithms are selected. In addition, it controls the level of outputs generated for each optimization cycle.

Q	A Optimiz	zation Parameters				
	General	Levenberg-Marquardt (LM)	Kuhn-Tucker (KT)	Default Constraints	Glass Polygon	Global Opt.
	Nur	min mber of Iterations	max 15	Optimization Ray Grid (ORGR) 16 x 16 ▼		
	We	ight on Aperture (WTA)	0.0000			
		Use Levenberg-Marquardt ( Use Kuhn-Tucker (KT)	LM)			
		Print detailed error function	t and iteration			
		Use real glasses instead of f	ictitious glasses using	g catalogue: Schott	<b>V</b>	
	Н	elp Apply	Close	Optimize	GO Te	erminate OPT

Figure 19.11: Optimization parameters main dialog.

The following commands allow control of the optimization process.

#### **19.15.1** Optimization Parameters for local Optimizers KT and LM

EDI OPT	Edit operating parameters for optimization algorithms. Note that the command 'EDI OPR' is obsolete but still supported. Instead, use of the 'EDI OPT' command is en- couraged.
MXC max_cycles	Maximum number of permitted cycles. The optimization will be terminated if that number of cycles is completed. Termination will probably occur before if the fractional improvement is less than the improvement factor (see IMPR command below).
MNC min_cycles	Minimum number of required cycles. Optimization will not exit earlier.

continued from previous page	
IMPR min_impr_factor	Fractional improvement. Optimization is terminated if the improvement of the error function is less than IMPR. Example: IMPR 0.01 corresponds to 1% improvement. Termination may occur before the maximum number of cycles (MXC) is reached.
ORGR num_opt_rays	Number of rays across pupil in optimization. Permissible values of num_opt_rays are 4, 8, 16, 32, 64, 128, 256 and 512. How- ever, ORGR must always be smaller than NRD. See the notes be- low.
OERR error_limit	Error limit. Optimization is terminated if the number of ray trace errors (if any) exceeds error_limit. Enter OERR 0 for disabling this feature.

#### Notes:

The optimization ray grid defines the number of rays across the pupil diameter during optimization. This setting must not be confused with the number of rays used for performance analysis (see NRD command). Setting the optimization ray grid (ORGR) to a value lower than NRD will only reduce the number of rays *during* optimization. For example, selecting ORGR 16x16 and NRD 32 will only use every second ray in the ray matrix during optimization. This accelerates the speed of optimization by a factor 4, whereas all performance analyses (e.g. spot, PSF, MTF, etc.) still use the 32x32 ray grid.

#### 19.15.2 Optimization Parameters for Global Optimizer GO

EDI OPT	Open dialog for editing operating parameters, provides several tabs for each optimization method (KT, LM, GO). For the global optimization see also Fig. 19.12.
GOH height	Global Optimization: Height of escape function.
GOW width	Global Optimization: Width of escape function.
GOT distance_tol	Global Optimization: Distance tolerance of escape function. De- fines the minimum distance in the parameter space from the pre- vious solution to constitute a new solution.
GOMXS max_solutions	Global Optimization: Maximum solutions.
GOV	Global optimization viewer. Invokes a dialog box for browsing through the different GO solutions and view their optical layout.
GOPT	Run (execute) the global optimization

#### Notes:

• If a solution is found in the global optimization (GO) process, it will be stored in the directory c:\programdata\optalix\gopt\. This is a fixed directory and cannot be changed. The

¢	* Optimization Parameters
	General Levenberg-Marquardt (LM) Kuhn-Tucker (KT) Default Constraints Glass Polygon Global Opt.
	Set parameters for global optimization using the escape function proposed by Isshiki.
	EscFkn HEIGHT 0.00000 Set default
	EscFkn WIDTH 1.00000
	EscFkn DISTANCE 1.00000 minimum value to constitute a new solution
	Max. Solutions
	File name prefix gopt
	Help Apply Close Optimize GO Terminate OPT

Figure 19.12: Global optimization parameters subdialog.

file name for this solution is constructed by the components file prefix, current number of the solution and the merit function value. All components are separated by an underscore "\_". Example: prefix\_number\_meritfkn.otx

• The button "Terminate OPT" in the lower right of the optimization parameter dialog (see Fig. 19.12) allows to stop a current optimization process, for example when an optimization takes too long or ist not converging, respectively for other reasons. This button works in all optimization options (KT, LM, GO). It is advisable to keep this (modeless) dialog (and the button) visible and not let is obscured by other dialogs or windows to ensure rapid access to this button.

## **19.16** Global Optimization: A worked Example

This section explains the parameter settings and steps needed to perform a global optimization. It is shown on the example global\_opt\_45-64\_Projection-lens.otx found in the examples library under optimization. A prerequisite of the global optimization is a working *local* optimization with well defined variables and constraints (merit function). The local optimization must converge and does not generate (raytrace) errors. The parameters in this example are already properly preset. The lens should be stored before a global search is started.

Make sure that a sufficient number of optimization variables are defined so that the design can "float" or "breathe". First, we test the local optimization using the KT method, where the output should be as follows (default constraints ignored):

Min.	Equal.	Inequal.	DampingF.	Improv.
0.421598	0.001380	1.527570	1.000000	
0.422651	0.005771	1.081881	0.1100528E-01	-0.00250
0.450504	0.040067	0.011254	0.2751319E-02	-0.06590
0.393552	0.094793	0.637684	0.2452433E-02	0.12642
0.397217	0.080271	0.361279	0.6131082E-03	-0.00931
0.400078	0.101365	0.188870	0.2452433E-02	-0.00720
0.388519	0.067179	0.244764	0.9809732E-02	0.02889
0.388303	0.046970	0.055582	0.3923893E-01	0.00056
	Min. 0.421598 0.422651 0.450504 0.393552 0.397217 0.400078 0.388519 0.388303	Min.Equal.0.4215980.0013800.4226510.0057710.4505040.0400670.3935520.0947930.3972170.0802710.4000780.1013650.3885190.0671790.3883030.046970	Min.Equal.Inequal.0.4215980.0013801.5275700.4226510.0057711.0818810.4505040.0400670.0112540.3935520.0947930.6376840.3972170.0802710.3612790.4000780.1013650.1888700.3885190.0671790.2447640.3883030.0469700.055582	Min.Equal.Inequal.DampingF.0.4215980.0013801.5275701.0000000.4226510.0057711.0818810.1100528E-010.4505040.0400670.0112540.2751319E-020.3935520.0947930.6376840.2452433E-020.3972170.0802710.3612790.6131082E-030.4000780.1013650.1888700.2452433E-020.3885190.0671790.2447640.9809732E-020.3883030.0469700.0555820.3923893E-01

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Ray errors encountered :	0				
Optimization stopped. Improvement	is less than	0.00100 (0.10%)			
Targets/Constraints	Target	Function	Error	Violation	
efl = 75	75.000000	74.998110	-0.001890		
spd 0	0.00000	0.009413	0.009413		

We see that the merit function converges and there are no errors. The parameters for the global optimization are edited by the optimization parameter dialog, invoked by the command EDI OPT or from the main menue *Optimization* -- > *Parameters Editor*. The last tab of this dialog, named "Global Opt." and shown in Fig. 19.12, allows editing of the main parameters H and W as well as the escape distance tolerance T of the parameter  $D_E$  (see eq. 19.7 and 19.8). This dialog is modeless, so it can (should) stay opened to allow always immediate access to edit the parameters or terminate the optimization.

The problem in the Isshiki escape function method is that the appropriate initial values for H, W and T are not known when starting the global optimization. The following empirical rules, as already mentioned in sect. 19.3 above, shall be repeated here to help in setting reasonable start values:

- The initial value of H shall be approximately the size of the error function that was obtained in the local optimization. The program first calculates the merit function from the local optimization and then sets H = meritfkn. This is the start value for H in the global optimization.
- The initial value of W can be safely set to 1.
- A distance threshold in the range 0.1 < T < 10 is advised. Low values of T create more solutions of similar shape, high values of T create fewer, but more independent solutions
- The merit function and its constraints must be well defined so that the local optimization safely converges, i.e. the local optimizer must not diverge, must not lead to infeasible solutions or violate optical laws. It is advisable that the optical system is locally optimized first. The parameters and constraints of your merit function will then also used in the global optimization.

Appropriate values for the parameters H, W and T are already preset in the example design. The global optimization is then started by the command GOPT, or from the main menue *Optimization* --> *Global Optimization*, or from the optimization parameter dialog shown in Fig. 19.12. The partial output from a global optimization run is:

• • •					
Searching no.:	2 MeritFkn =	0.3788	Escape_dist	= 3.4114	
Adapting ecape	function W,H:	1.092	0.845		
Searching no.:	3 MeritFkn =	0.3800	Escape_dist	= 0.0036	
Adapting ecape	function W,H:	1.190	1.099		
Searching no.:	4 MeritFkn =	0.3763	Escape_dist	= 6.8225	
Solution found:	1 MeritFkn =	0.3763	C:\ProgramD	ata\OpTaliX\gopt	\GOPT_1_0.3763.otx
Searching no.:	1 MeritFkn =	0.3773	Escape_dist	= 0.6472	
Adapting ecape	function W,H:	1.226	1.428		
Searching no.:	2 MeritFkn =	0.3800	Escape_dist	= 1.7965	

The program constantly does a local optimization with and without the escape function applied (the searching modus) and tests constantly if the parameter change (the escape distance) exceeds the predefined escape tolerance T. If the escape distance did not meet the escape tolerance, i.e. the escape from the local minimum failed, the parameter H and W are successively increased by small amounts until the escape tolerance T is reached. In case this escape condition is fulfilled, a new solution is filed. At the end of the global optimization run, either when the maximum number of solutions is reached or if the process was interrupted by pressing the "Terminate OPT" button, the solutions can be found in the directory c:\programdata\optalix\gopt\. The global solutions can be conveniently browsed by the global solutions viewer, command GOV, see also Fig. 19.13.



Figure 19.13: Global optimization viewer. Browse conveniently through all solutions from a global optimization run.



Figure 19.14: Solutions from a global optimization search. The upper left design is the start design.

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# Coatings

Optical components are usually coated with thin layers of solid materials for the purpose of altering their physical or optical properties. Depending on the application, only one thin layer or a stack of as many as fifty to over hundred layers are deposited to produce the desired optical behaviour. The terms "*multi-layer*" respectively "*coating*" in the following sections are used as generic terms for single or multiple thin films on optical surfaces.

The design, analysis and optimization of multi-layer coatings (thin films) is seamlessly integrated to OpTaliX. Thus, it is not necessary to perform a multi-layer design in a separate program and then laboriously transfer (import) the data to OpTaliX.

One single coating can be loaded during a session. It will be stored in memory in parallel to the classical optical surface data and it can be modified, optimized and analyzed independently from the optical system. Once the performance is considered sufficient, it may be attached to a particular optical surface or a range of surfaces (see also section 20.5).

OpTaliX also allows access to coating designs from other thin-film packages such as "The Essential MacLeod" and "Thin-Film-Calc (TFCalc)". See sect. 29 (page 491) on importing coating designs from these packages.

**Nomenclature:** In the commands and the options to follow, "COA" always refers to the single coating stored in the coating editor; it can be independently edited and optimized from the system prescription data. If "MUL" is indicated in a command syntax, it refers to the coating *attached to a surface*. Note that a coating attached to a surface cannot be modified, it can only be removed (DEL MUL) or overwritten (ATT COA) by another coating stored in a file or in the coating editor.

## 20.1 Editing Coating Data

Coating prescriptions may be edited either from the command line (sect. 6) or from the GUI via a spreadsheet editor giving access to all layer parameters. The coating editor is invoked by the command EDI COA

Note that the coating editor only allows modification of layer data (layer material, layer thickness, etc.) of a coating stack. The conditions of use of the coating stack (e.g. incidence angle, plotting parameters) are defined in the coating configuration dialog.

## **20.2** Coating Configuration

The coating configuration data pertain to the use of thin-film multilayer coatings. For example, coating configuration data are reference wavelength, incident angle, plot or analysis wavelength, etc. A

	MATERIAL	Pick	Index (real)	Index (imag.)	OTH	PTH (micron)	Pick	P-Factor	Var	
1		0	1.000000	0.000000	0.000000	0.000000	0	1.0000		Γ
2		0	1.380000	0.000000	0.300300	0.110981	0	1.0000		
3		0	2.250000	0.000000	0.128100	0.029036	0	1.0000		
4		0	1.380000	0.000000	0.065700	0.024280	0	1.0000		
5		0	2.250000	0.000000	0.678900	0.153884	0	1.0000		
6		0	1.380000	0.000000	0.071800	0.026535	0	1.0000		
7		0	2.250000	0.000000	0.084000	0.019040	0	1.0000		
8		0	1.520000	0.000000	0.000000	0.000000	0	1.0000		

Figure 20.1: Coating editor, invoked by the command EDI COA.

dialog box for editing coating configuration data is invoked by the EDI CCFG command (see also command description in next section).

**Important note:** In this context, coating configuration data must not be confused with **system** configuration data (see EDI CNF command).

# 20.3 Coating Command Line:

EDI CCFG	Coating configuration dialog
	Coating configuration dialog.
RES COA [coating_name]	Restore a coating from file and keep it in memory (in parallel to the lens data). The standard file extension is ".otc". In absence of the extension, it will be automatically added. If the optional parameter coating_name is missing, a dialog box will be opened. Once loaded into memory, the coating may be attached to an optical surface using the ATT command (see be- low). The file specified by coating_name must reside in the coating directory which is by default \$i\coatings. Thus, it is not required to specify this path information explicitly. Ex- amples of valid coating-file commands are: res coa ar_coat.otc res coa ar_coat
SAV COA [coating_name]	Save a coating to file "coating_name". The default directory
	where to the coating prescription is saved is \$i\coatings.
	Do not modify this setting, because the stored file may not be
	loaded later $(OpTaliX$ expects all coating files in this direc-
	tory). In absence of coating_name, a dialog box is opened.
LIS MUL [sk sij]	Lists multilayer coatings attached to surfaces.
DEL MUL [sk si,,j]	Delete multilayer coating on surfaces sk sij. The surface is then assumed uncoated. In subsequent polarization and transmission analyses, Fresnel equations are used.
EDI COA	Edit coating data using a spreadsheet.
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INV COA	Invert a multilayer coating, including the incident/substrate me- dia.
CREF	Reference wavelength in $\mu$ m of thin-film multilayer coating
coating_wavelength	stack. The coating must have been loaded before (see RES COA command).
OTH lij	Optical thickness (in wavelength units defined by the base
layer_thickness	wavelength). The physical thickness will be automatically eval- uated according to the base wavelength.
PTH lij phys_thick	Physical thickness (in mm) of the layer(s) lk lij. The optical thickness will be automatically evaluated according to
	the base wavelength.
INS lij	Insert layer i to j
DEL lij	Delete layer i to j
GLA lij material	Material (glass) for layers i to j.
IND lij real_index	Complex index of refraction of layer(s) i to j. Takes only ef-
imag_index	fect, if no layer material (see GLA command above) is specified.
ATT sk sij [ FILE coating_name   DEF ]	Attach a multi-layer coating, stored in memory or in a file to surface(s) $sk sij$ . The coating name refers to a file containing the coating prescription. The coating file MUST reside in the standard coating directory $OpTaliX$ (usually $i\coatings$ ). If the option [FILE coating_name] is absent, the actual coating stored in memory will be attached.
	The optional parameter DEF assigns a 'default' coating, con- sisting of single quarter-wave thickness MgF2 layer to the des- ignated surfaces.
MAN [ R   T   A ]	Numerical analysis of multi-layer performance. The analysis may be performed for : R = reflection, T = transmission. A = absorption
[ANG incid_angle]	(transmission, reflection, absorption) will be printed. An incidence angle (in degrees) can be optionally provided. In this case the ANG qualifier is obligatory. If ANG is omitted, the incidence angle specified in the coating configuration dialog (see EDI CCFG) is used.
COA LAM R T RP TP	<ul> <li>Plot reflection/transmission properties vs. wavelength (LAM = λ).</li> <li>R = reflection</li> <li>T = transmission</li> <li>RP = phase change on reflection</li> <li>TP = phase change on transmission</li> </ul>
	continued on next page

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COA FLD R T	Plot reflection/transmission properties vs. field (i.e. incidence angle). The wavelength used is the coating reference wave- length, which must not be confused with the reference wave- length in the optical system (see REF command). R = reflection T = transmission
COA FLA R T	Plot reflection/transmission properties vs. field (i.e. incidence angle) and wavelength as 2-dimensional surface plot. R = reflection T = transmission
COA GD R T	Plot group delay vs. wavelength. R = reflection T = transmission
COA GDD R T	Plot group delay dispersion (or group velocity dispersion) vs. wavelength. R = reflection T = transmission
FTAR	Define performance targets (see section 20.9.2 on page 397).
F.O.B.I.	Run the coating optimization.
	Selects the colour list used for coating analysis plots correspond- ing to S, T and A (average). With no colours specified, colours are set to default settings. Examples: cls coa red gre blu! defines red, green and blue for S, T and average plane. cls coa! no colours specified, default coating colours are se- lected. See also names of predefined colours and their definition in sect. 28.1, page 489.
EXP COA R T plane [fil filename]	<pre>Save (export) coating reflection/transmission performance to a file in ASCII format. R T specifies reflection/transmission plane = polarization plane, S = s-plane, P = p-plane, A = aver- age plane (S+P)/2 By default, output is directed to the text output screen. If a file name is specified ('fil' option), output is written to a file des- ignated by 'filename'. This export option uses the parameters (max. angle, wavelength range, etc.) set in the general coating configuration (see also EDI CCFG command) Example: exp coa R A fil c:\mycoat.txt: exports reflection properties (R) for average polarization (A) to file c:\mycoat.txt.</pre>

## **Spreadsheet Entry:**

The spreadsheet is invoked by the command EDI COA or from the main menu Coatings  $\rightarrow$  Edit Layers.

📢 E:\opx4\Coatings\dwdm_1.otc						×		
	MATERIAL	Index (real)	Index (imag.)	OTH	PTH (micron)	P-Factor	Var	•
1		1.000000	0.000000	0.000000	0.000000	0.0000		
2	SI02	1.444018	0.000000	0.250000	0.268348	0.0000	N	
3	TA205	1.997176	0.000091	0.250000	0.194024	0.0000	N	
4	SI02	1.444018	0.000000	0.250000	0.268348	0.0000	N	
5	TA205	1.997176	0.000091	0.250000	0.194024	0.0000		
6	SI02	1.444018	0.000000	0.250000	0.268348	0.0000		
7	TA205	1.997176	0.000091	0.250000	0.194024	0.0000		
8	SI02	1.444018	0.000000	0.250000	0.268348	0.0000		
9	TA205	1.997176	0.000091	0.250000	0.194024	0.0000		
10	SI02	1.444018	0.000000	0.250000	0.268348	0.0000		
11	TA205	1.997176	0.000091	0.250000	0.194024	0.0000		
12	SI02	1.444018	0.000000	0.250000	0.268348	0.0000		
13	TA205	1.997176	0.000091	0.250000	0.194024	0.0000		-
	Insert [	Delete			Close			

Figure 20.2: Editing coating data using a spreadsheet.

The meaning of the columns is:

Material	The material can be any glass/material name from the glass catalogue. If a blank name is specified, the complex index of refraction must be entered, which is always referred to the reference wavelength. This index is used for all wavelengths, hence material dispersion cannot be accounted for. For catalog glasses (i.e. a material name is given), dispersion will always be taken into account. New materials can be defined by the user with the material editor (see sect. $20.10$ ).
Index (real)	The real part $n$ of the complex index of refraction, which is defined as $(n - ik)$ .
Index (imag.)	The imaginary part $k$ of the complex index of refraction $(n - ik)$ , also known as extinction coefficient.
ОТН	The optical thickness. It is the physical thickness PTH (as it would be measured by a ruler) multiplied by the refractive index of the material and divided by the reference wavelength, i.e. $OTH = n \cdot PTH/\lambda_0$ . For example, 0.25 would be a quarter-wave layer, i.e. the optical path is exactly one quarter of a wave.
РТН	The physical thickness as it would be measured by a ruler. The numbers in the column are always in microns.
P-Factor	The P-factor describes the packing density, since materials in thin films seldom have bulk properties. Thin films usually exhibit a pronounced columnar morphology with pore-shaped voids between the columns. This reduces film packing density and in turn its optical properties. The P-factor is between 0 and 1. When P is 1, the whole void space is occupied by the material, this is equivalent to a bulk material. To model varying packing density, the refractive index of the layer is given by $n = (1 - P) [(1 - f) + fn_{\nu}] + Pn_s$
Var	A layer thickness can be made variable by checking the appropriate box. Variable layer thicknesses are required for coating optimization (refinement).

## 20.4 Composing a new Coating

New coating designs can be created using a shorthand notation on the basis of quarter-wave layers. This option requires specification of two different materials, which are represented by capital letters (symbols) such as **H**, **L**, **A**, **B**, etc. Commonly, the symbol H is used to represent a high-index material and L for a low-index material. The symbols can be combined into a formula using a sequence, such as HLHL or AH2LHB. The incident medium is assumed to be left of the formula and the substrate to the right. Air and substrate are always added to the stack and need not be specified in the formula.

Layer thicknesses other than quarter-wave are represented by multiples of the basic units. For example, 2.5H is 2.5\*0.25 waves = 0.625 full waves. Repeated sequences can be included in brackets with an exponent or replication factor. Exponentiation is indicated by the caret symbol  $^{\circ}$  or alternatively by the asterisk symbol \*, e.g. (HL) $^{\circ}$ 6 or (HL)\*6. The formula is then interpreted and expanded into a sequence of layers. The following table gives examples of valid and invalid shorthand notations:

correct	invalid	Remarks to the invalid form
HL	(HL)	Brackets always require an exponent
2HL	(H^2L)	Exponent not allowed within brackets.
(HL)^2	(HL) ^	Exponent number missing
(HL)^2 L(HL)^3	(HL)^2L(HL)^3	Blank space after exponent is missing

Note the space following the exponent, which is required. If it is omitted, the formula will be rejected. Nesting of brackets is NOT permitted. Air and substrate need not necessarily be specified, as they are always automatically created.

#### **Dialog based entry:**

A dialog box is invoked from the menu *Coatings*  $\rightarrow$  *Compose new coating*. It allows entry of the material symbols and the corresponding materials, which are chosen from dropdown lists. Since each symbol represents an optical thickness of a quarter-wave, there is no option for thickness entry. Once the symbols have been defined the shorthand notation can be entered in the corresponding string field. In the example below, three materials are defined, which are represented by the symbols H, L and B.

📢 Coating Generator				
Creates a coating design already loaded coating w	using shortha ill be overwritt	nd notation on the basi en. Materials are repres	is of quarter-wa ented by letter	ave layers. An r symbols.
	SYMBOL	Material		
	Н	TA205	-	
	L	SI02	-	
	В	PBF2	<b>•</b> •	
	4		Þ	
Shorthand notation:	L(HL)^6 (LBI	H)^2		
	Example: L(0	).5HL)^2 H (LH)^4 H		
Help Co	onfig.	C	ancel	ОК

Figure 20.3: Dialog box to defining a new coating stack. Symbols (e.g. H or L) must first be assigned to materials, which can then be used in the shorthand notation, e.g.  $L(HL)^{-6}$ .

#### **Command Line Entry:**

FCOMP 'formula'	Film compose. Creates a new quarter-wave coating stack, which is described by a formula. Since the formula may contain blanks, it must be enclosed in quotation marks.					
	Example: fcomp 'L(HL)^3 B(HL)^6'					
	Assign a symbol to a material. For example,					
	FMAT H TIO2 assigns the symbol "H" to the material					
FSYM symbol material	"TiO2".					
	This makes the symbol "H" available to defining a coating					
	formula using the command FCOMP (see above).					

## 20.5 Specifying Coatings on Surfaces (Coating Attachment)

There are two methods to specifying coatings on optical surfaces:

- 1. Assign a coating, which is stored in a file, directly. This means specifying a coating name.
- 2. Load a coating into the coating editor and then view, analyse or optimize it. Once the performance is considered sufficient, attach it to a lens surface using the ATT command. Attach a 'default' coating (single quarter wave  $M_gF_2$  layer) to optical surfaces by the "ATT sk—si..j DEF" command (see also comments below).

By default, air-glass surfaces are assumed uncoated. On reflecting surfaces (mirrors, see REFL) and total reflecting (TIR) surfaces 100% reflectivity will be assumed.

## **20.5.1** Default (Single Layer $M_gF_2$ ) Coating

In addition to user-defined coatings a 'default' coating may be assigned to optical interfaces in absence of any other information. A default coating consists of a single layer quarter wave  $M_gF_2$  layer centered at the reference wavelength (see also section 17.1).

In the command line, a single layer  $(M_gF_2)$  coating is defined (i.e. attached to a surface) by ATT sk|si..j DEF

In the surface editor, enter "DEFCOAT" in the column labelled "Coating" (see Fig. 20.4).

													]	De on	efines a sing surfaces 1	le l - 2	MgF <sub>2</sub>	laye
<mark>ریھ</mark> 5u	rface Edi	itor: E:\optalix\e	kam	ples\Misc\D0	DUBLE	_GAUSS.OTX											_	
Stand	dard Data	Decenter, Tilts A	sph	ere GRIN S	olves	Special Aperture	s	Hologram 🗍	vlis	c.								
	TYPE	Radius		Distance		GLASS		APE-Y	×.	Shape		Glb	THR		Comment		oating	
OBJ	S	0.0000000		0.1000000E+2	21			0.00	0	circular 📘	-	0	0.00000					
1	S	28.7248827		4.37332	29	BSM24		15.00	1	circular 🗖	-	0	0.00000			DEF	COAT	
2	S	94.2300334		0.149090	)8			14.60	0	circular 💽	-	0	0.00000			DEF	COAT	7-1
3	S	17.4436362		6.21211	5	SK1		12.71	0	circular 💽	-	0	0.00000					
4	S	0.0000000		1.88848	33	F15		12.26	0	circular 💽	-	0	0.00000					
5	S	10.7346033		7,55393	12			8.48	0	circular 📘	-	0	0.00000					
4	10	0.0000000		0 (0000				1			-		0 00000			1		
EFL = MAG	50.00024 = 0.00000	BFL = 31.9 0 SYL = 37.9	5689 5211	3 EPD 7 OAL	= 25.0 = 69.0	00000 🔽	PIM	1										
Pos.	1 🔻	Insert Surf. Inse	ert Fi	le 🛛 Delete Sur	f.	Help Clos	se											

Figure 20.4: Defining 'default' coatings (i.e. single quarter wave layer  $M_g F_2$ ) in the surface editor.

See also section 8.36.1 for more details.

## 20.6 Phase Changes introduced by Coatings

The phase change that occurs at a coating when polarization ray tracing is active (POL YES) is automatically considered in the optical path length. That is, the optical path difference introduced by the finite thickness of a coating attached to a surface is added to the optical path length (OPL). This may result in different optical path difference (OPD) and correspondingly different diffraction analysis results (MTF, PSF, etc), depending on whether coatings are attached to surfaces or not.

Phase changes that occur on coatings can normally be neglected, however, on high numerical aperture systems or wide-angle systems with steep incidence angles on optical surfaces coatings may have a noticeable effect on phase (=wavefront) response.

## 20.7 Coating Thickness Variation

Usually it is assumed that thicknesses of layers in thin film stack is uniform over the whole area of the lens surface. In practice, however, there may be special conditions for which this assumption is not valid. For example, steep curved surfaces are very hard to coat uniformly. Due to the deposition process the overall thickness of the coating stack at curved surfaces gets thinner in the outer zones of the lens surface. It is obvious, that the performance (reflectivity, transmissivity, phase) of the coating will be different at the surface vertex (where rays usually hit the surface at near normal incidence) compared to the rim of the lens.

The most prominent effect of coating thickness variations are seen on transmissivity and reflectivity. However, phase effects induced by variations of coating thickness may affect the overall performane of a system, e.g. in systems with strongly curved surfaces, wide angles, or diffraction limited systems.

In order to model this effect, the thickness profile of a coating can be specified by polynomial functions. Two forms are available:

- Radial thickness variation, i.e. coating thickness variation exhibits rotational symmetry,
- Non-rotational symmetry of coating thickness over surface.

**Hint:** Use the commands "POL Y" and "TRA Y" (without the quotes) to include variations of coating thicknesses in analyses, such as wavefront, PSF, MTF, etc.

#### 20.7.1 Radial Thickness Variation

The overall coating thickness is described as a function of the radial coordinate on a surface by

$$s_c = a_1 + a_2 r^2 + a_3 r^4 + a_4 r^6 + a_5 r^8$$
(20.1)

where  $s_c$  is the scaling factor for the nominal coating thickness and  $r = \sqrt{x^2 + y^2}$  is the radial coordinate measured from the surface vertex. All layers of a given coating stack will be scaled by  $s_c$ . The scaling factor  $s_c$  is expected to be a number between 0 and 1. Negative values of  $s_c$  are not allowed, respectively are set to  $s_c = 0$  in the analysis. The coefficients  $a_i$  are specified by the command

CTV NO|RAD|XY sk|si..j ck|ci..j coeff\_1 coeff\_2 ...

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	Coating thickness variation defined by either radial (RAD) or non-						
	symmetrical (XY) polynomial. Enter the coefficients coeff_1,						
	coeff_2, etc, as given in Eq. 20.1. Coating thickness variation						
	is removed from a surface if $C1 = 1$ and all other coefficients are						
	zero.						
	Examples:						
	ctv rad s3 c2 -0.002						
	ctv rad s3 c25 0.01 0.02 0.03						
	ctv xy s23 c4 -0.002						
	See also sect. 20.7.2 for a description of the non-symmetrical						
	(XY) coating thickness variation.						
EDI CTV	Edit coefficients of coating thickness variation in a spreadsheet						
	editor.						
	Plot coating thickness variation (CTV) for a given surface sk.						
	Plots can be made in various styles specified by the optional pa-						
	rameter style:						
	WIR : wire-frame.						
PLO CTV sk [style]	CON : contour plot,						
	FAL : false colour plot,						
	XY : slices in X- and Y-direction.						
	The default plot style is wireframe.						
	Activate/deactivate polarization analysis. Turn on polarization						
POL Y N]	analysis (pol v) if you want to analyze the effects of coating						
	thickness variation on wavefront.						

See also related commands:

LIS MUL	List multilayer coatings attached to optical surfaces,
PMA	Plot system pupil map (i.e. transmission in system exit pupil).
POL Y	Turn on polarization analysis to see CTV effects on wavefront.

#### **Example:**

We assume a decrease of the coating thickness by a radial quadratic function. The thickness of the coating stack at the rim of a lens reduces to 70% of the thickness at its vertex, i.e. the thickness scaling factor at the rim is 0.7. From Eq. 20.1 we have

$$0.7 = a_1 + a_2 r^2$$

Assuming furthermore a lens diameter of 50 mm (r = 25mm), we obtain

$$0.7 = a_1 + a_2 \cdot 25^2$$

Since the thickness scaling factor s - c must be 1 at r = 0 (vertex),  $a_1$  must be 1. Then,  $a_2$  is calculated by

$$a_2 = \frac{s_c - 1}{r^2} = \frac{0.7 - 1}{25^2} = -0.00048$$

The commands for this example are then (assuming coating thickness variation at surface 3)

395
```
ctv s3 c1 1 ! a_1 = 1
ctv s3 c2 -0.00048 ! a_2 = -0.00048
```

#### 20.7.2 Non-symmetrical Thickness Variation

Almost arbitrary (non-symmetrical) coating thickness variations can be modeled by a 2-dimensional polynomial of the form

$$s_{c} = a_{1} + a_{2}x + a_{3}x^{2} + a_{4}x^{3} + a_{5}y + a_{6}y^{2} + a_{7}y^{3} + a_{8}xy + a_{9}x^{2}y + a_{10}xy^{2}$$
(20.2)

where  $s_c$  is the scaling factor for the nominal coating thickness and x, y are the physical coordinates on the surface measured from the surface vertex. All layers of a given coating stack will be scaled by  $s_c$ . The coefficients  $a_1$  to  $a_{10}$  are specified by the CTV command as given in the previous section 20.7.1, (page 394).

The coating thickness variation on specific surfaces can be plotted by the command PLO CTV. Set POL Y to see effects of coating thickness variation (CTV) on wavefront.

## 20.8 Accounting for the Phase in an Optical Coating

The wavefront in an optical system may be distorted by optical coatings, depending on the type of coating, the incidence angle and the wavelength. Optical coatings introduce additional phase effects in an optical system, and therefore may have a significant impact on the wavefront passing through an optical system, in particular if the thicknesses of the coating layers are not uniform over the area of deposition.

Unfortunately, there is no commonly accepted method to which surface the phase is referred to, it can be the incident surface of a coating or to the exiting surface of a coating. Depending on the definition, the geometrical thickness of a coating stack must be included or not in order to obtain a correct phase/wavefront representation.

In general, the phase introduced by an optical coating is expressed by

$$\Phi_{wf} = \Phi + \frac{2\pi n_0 \cdot d \cdot \cos(\theta_0)}{\lambda}$$
(20.3)

where  $\Phi$  is the phase as usually calculated by thin film codes,  $n_0$  is the refractive index of the entrance medium, d is the total thickness of the coating,  $\theta_0$  is the angle of incidence on the coating.

OpTaliX uses the convention defined in the MacLeod package where the geometrical term (i.e. the right term) in eq. 20.3 is already included in the phase result. Other thin film packages may use different definitions that must be carefully checked.

## **20.9** Thin Film Optimization (Refinement)

Optimization is a process for the improvement of design performance. It requires an already existing starting design. Optimization does not synthesize a coating design as it would be possible by other methods (e.g. building a system virtually from scratch by automatically adding layers, such as the so-called "Needle" method, simulated annealing or "Optimac").

### 20.9.1 Variables

Variables are thicknesses of layers. They can be defined in the coating spreadsheet editor. If the appropriate box is checked, the layer thickness is variable during optimization, if it is unchecked, the thickness will not be changed in the optimization. See also page 391 for editing coating data.

### 20.9.2 Targets

Optimization (refinement) of coatings requires first of all the definition of a target performance. The actual performance is compared with the targets and the deviation of actual and required performance is expressed by the function of merit.

In coating optimization, targets are a series of reflectance or transmittance values at discrete wavelengths. Since there may be many targets required in complex designs, a dialog box supports the definition of targets. It is called from the main menu selecting *Coatings* -> *Targets*.



Figure 20.5: Targets dialog box.

Targets are created by specifying a wavelength range and the number of wavelengths in that range. The target values in this range may be between 0 and 1, corresponding to 0% or 100% transmittance or reflectance, respectively. Targets can be referred to the S-plane, P-plane or an average value between S- and P-plane by selecting the appropriate radio buttons, as shown below:



**Weights** are usually set to 1, but they may be between 0 and 100. A weight 0 means, that this performance target does not contribute to the merit function. The higher a weight is, the more will the aberration (difference of actual performance from target) contribute to the merit function.

Pressing the **Add** button will create the targets. Several wavelength ranges with different targets (reflection, transmission, S- P- or average plane) can be combined to define more complex performance constraints.

**Clear all**: Pressing this button will clear all targets.

**Deleting targets**: Individual targets can be deleted by selecting a group of rows in the targets table. For example, deleting the variables (rows) numbered 2 to 3 is accomplished first by clicking onto the row label 2 (the whole row is marked), then holding the shift key and clicking onto row label 3. Rows 2 and 3 are now marked black. Pressing the **Del** button on the keyboard will delete the rows. Alternatively, **Ctrl-X** will also delete the rows and the contents of the deleted rows is additionally copied to the clipboard.

## 20.9.3 Run Coating Optimization

Having defined variables and performance targets, the coating can now be optimized (refined). This is accomplished in the command line by typing FOPT or from the main menu selecting *Coatings*  $\rightarrow$  *Optimize coating*.

	Thin film optimization, requires proper setting of targets and vari-
EODT [n it on]	ables. The optimization stops after n_iter cycles, independent
FOPI [n_iter]	whether a local minimum has been reached. If n_iter is omitted,
	optimization stops at the apparent (local) minimum.

## 20.10 Coating Material Editor

The coating material editor manages a database of materials used in thin-films. OpTaliX provides a library of predefined coating materials (which cannot be modified) and a library of private (i.e. user-defined) coating materials which can be modified (editing, adding new materials or deleting unnecessary materials).

Thin film materials are both dispersive and absorbing. This is the major distinction from "conventional" glasses used in ray tracing which are only modelled by their dispersive properties. "Conventional" glasses, like BK7, exhibit almost negligible absorption within the wavelength range for which dispersion coefficients are valid.

Unlike "conventional" glasses, thin-film materials are defined by the refractive index n and the extinction coefficient k (i.e. the imaginary part of the complex index of refraction) against wavelength  $\lambda$  (given in microns).

If necessary, the values are interpolated or extrapolated. Interpolation is linear. Extrapolation keeps the last value from the material table. A linear interpolation is used for calculating (n, k) pairs rather than dispersive formulae because of the wide range of different materials and conditions that are involved. Metals, for example, cannot be represented by the common normal dispersion formulae (such as Sellmeier or Herzberger equations) that are useful only for non-absorbing (dielectric) materials over a limited spectral region.

Private thin-film materials can be edited in the coating material editor which is invoked from the main menu by selecting *Coatings* --> *Material Editor* or from the command line by

EDI CMAT	Edit coating (thin-film) materials. This command opens a dialog box as
	shown in Fig. 20.6. Each material can be defined by up to $100 (n, k)$ pairs.
	The wavelengths do not need to be equally spaced.

Material Editor Private Materials Catalogue Mate	rials				×
Select Material	Materi SiO2,	al description (up test example	o to 200 charact	ters)	
Navy Material		Wavelength	Index (real)	Index (imag)	
New Material	1	0.21440	1.53371	0.00000	
Delete Material	2	0.26500	1.50004	0.00000	
	3	0.30200	1.48719	0.00000	
	4	0.40400	1.46961	0.00000	
	5	0.50800	1.46187	0.00000	
	6	0.58900	1.45841	0.00000	
	7	0.65600	1.45637	0.00000	
	-	0.05200	1.45040	0.00000	
Help		Cancel	OK		

Figure 20.6: Editor for defining coating materials.

## 20.11 Coating Index Profile

Produces a plot of refractive index against thickness. In the index profile, the incident medium (typically Air) is on the left and the emergent medium, or substrate, on the right.



Figure 20.7: Coating Index Profile

Refractive index profiles can be shown by real part, imaginary part or both components simultaneously.

## 20.12 Export Coating Performance Data

The performance of optical coatings (reflection, transmission, phase) can be exported to an Excel spreadsheet. From the command line, this is accomplished by the command

	Perform multilayer analysis and export the transmis- sion/reflection/phase performance to an Excel spreadsheet.
MAN R T XLS file_name	Example: man r xls c:\temp\refl.xls

From the menu, select *Coatings / Reflection / Numeric, as Excel file* (see Fig. 20.8):



Figure 20.8: Menu for exporting coating performance to Excel.

## 20.13 Basic Relations

Generally, a thin film coating is a media, whose properties are constant throughout each plane perpendicular to a fixed direction and is called a *stratified medium*. The calculation scheme presented in this section follows the treatment by Macleod [32]. A similar treatment is found in Born and Wolf [4].

The electric field E and the magnetic field H at one boundary of a film are related to the fields E' and H' at the other boundary by two linear simultaneous algebraic equations, written in matrix form:

$$\left(\begin{array}{c}E\\H\end{array}\right) = M_j \cdot \left(\begin{array}{c}E'\\H'\end{array}\right)$$
(20.4)

where the M is the characteristic matrix for an individual layer j:

$$M_j = \begin{bmatrix} \cos(\delta_j) & -\frac{i}{p_j}\sin(\delta_j) \\ -ip_j\sin(\delta_j) & \cos(\delta_j) \end{bmatrix} = \begin{bmatrix} m_{11} & m_{12} \\ m_{21} & m_{22} \end{bmatrix}$$
(20.5)

For a multi-layer stack containing m layers, the calculation of reflectance, transmission and phase properties involves successive multiplication of the characteristics matrix

$$\begin{bmatrix} B \\ C \end{bmatrix} = \left\{ \prod_{j=1}^{m} \begin{bmatrix} \cos(\delta_j) & -\frac{i}{p_j}\sin(\delta_j) \\ -ip_j\sin(\delta_j) & \cos(\delta_j) \end{bmatrix} \right\} \cdot \begin{bmatrix} 1 \\ p_{sub} \end{bmatrix}$$
(20.6)

with

 $k_0 = \frac{2\pi}{\lambda}$ 

 $N_j = n - ik$  = complex refractive index of layer *j*. *n* is the real refractive index and *k* is known as the extinction coefficient. *k* is related to the absorption coefficient  $\alpha$  by  $\alpha = 4\pi k/\lambda$ .

 $d_j$  = physical thickness of layer j

- $\theta_j$  = refraction angle at boundary of layer *j*, given by Snell's law:  $n_0 sin\theta_0 = n_j sin\theta_j$ , the subscript 0 denoting the incident medium.
- $\begin{array}{ll} \delta_j &= 2\pi N_j d_j cos \theta_j / \lambda \\ i &= \sqrt{-1} \end{array}$

We obtain different characteristic matrices for TE- and TM-waves<sup>1</sup>. For a TE wave we set  $p_j = N_j/\cos\theta_j$ . For a TM wave, the same equations hold, with  $p_j$  replaced by  $q_j = N_j \cdot \cos\theta_j$ . The reflection and transmission coefficients of the film are then obtained by:

$$r = \frac{m_{11}p_0 + m_{12}p_0p_{sub} - (m_{21} + m_{22}p_{sub})}{m_{11}p_0 + m_{12}p_0p_{sub} + (m_{21} + m_{22}p_{sub})} = \frac{p_0B - C}{p_0B + C}$$
(20.7)

$$t = \frac{2p_0}{m_{11}p_0 + m_{12}p_0p_{sub} + (m_{21} + m_{22}p_{sub})} = \frac{2p_0}{p_0B + C}$$
(20.8)

In terms of r and t, the *reflectivity* and *transmissivity* are:

$$\mathcal{R} = |r|^2 = \frac{(p_0 B - C)(p_0 B - C)^*}{(p_0 B + C)(p_0 B + C)^*}$$
(20.9)

$$\mathcal{T} = \frac{p_0}{p_{sub}} |t|^2 = \frac{4p_0 Real(p_{sub})}{(p_0 B + C)(p_0 B + C)^*}$$
(20.10)

The phase  $\phi_r$  of r may be called the *phase change on reflection* and the phase  $\phi_t$  of t the *phase change on transmission*. The phase change  $\phi_r$  is referred to the first surface of discontinuity, whilst the phase change  $\phi_t$  is referred to the plane boundary between the stratified medium and the last semi-infinite medium.

We have different phase changes for each plane of incidence (S and P) and we obtain for the phase changes on reflection and transmission:

$$\phi_r = \phi_{r(S-plane)} - \phi_{r(P-plane)}$$
  

$$\phi_t = \phi_{t(S-plane)} - \phi_{t(P-plane)}$$
(20.11)

 $n_1 = \sqrt{n_0 \cdot n_{sub}}$ 

When a layer is a quarter-wave thick, particularly simple results can be obtained. A few special cases are summarized here (with  $n_0$  = index of incident medium,  $n_s$  = index of substrate):

Single layer, zero reflectivity requires

Double quarter, single minimum, zero reflectivity requires  $\frac{n_2}{n_1} = \sqrt{\frac{n_{sub}}{n_0}}$ 

<sup>&</sup>lt;sup>1</sup>TE-wave = transverse electric wave: The electric vector is perpendicular to plane of incidence (S-plane, from German "senkrecht"). TM-wave = transverse magnetic wave: The magnetic vector is parallel to plane of incidence (P-plane, from German "parallel")

Double quarter, double minimum, zero reflectivity requires

 $n_1 \cdot n_2 = n_0 \cdot n_{sub}$ 

Triple Layer, Minimum reflectivity is accomplished for:

$$n_1 \cdot n_3 = n_0 \cdot n_{sub}$$
$$n_2^2 = n_0 \cdot n_{sub}$$

# **Environmental Analysis**

The environmental analysis takes into account the changes in lens data which result from changes in temperature and pressure. The changed system becomes the basis for all subsequent analyses, e.g. image evaluation. The changed system can be saved and also optimization can be performed to test active compensation schemes. The environmental parameters can be applied to the entire optical system or individual parts to model temperature and/or pressure gradients.

It is important to note the initial conditions for all lens data:

- The nominal temperature is  $20^{\circ}C$ ,
- all spaces, including the object and image space, are filled with air at sea level pressure  $(1013.25 \cdot 10^9 \text{ Pa})$ ,
- the index of air is regarded to be 1.0. This is also the assumption made in glass catalogues. See also section 13.8.

These conditions need not to be entered explicitly, they are assumed as default. When temperature and/or pressure is altered, all data are converted from relative indices to absolute indices, relative to vacuum as 1.0. This conversion is automatically done and does not require user interaction. If no other environmental changes are made to the optical system (i.e. it remains at 20°C, 760 mm Hg), the same optical answers are given before and after this process. The only difference is, that indices are now referred to vacuum. For example, the command TEM sa 20 assigns the temperature 20°C to all surfaces. This, however, is the initial default condition and the system must show the same optical performance. The surface listing (see LIS) then reports indices relative to vacuum. Air, for example, has an index of refraction of approximately 1.000273 in the visible spectrum. Air spaces will automatically be filled with the pre-stored "material" AIR to account for the (small) dispersion of air.

## 21.1 Temperature

A temperature distribution can be assigned to a range of surfaces or to the entire lens system.

	Temperature at surface(s) sij. The system data are changed immediately! Temperature gradients
	can be modelled by assigning different temperatures
TEM sij sa temperature	to individual surface ranges sij.
	Example:
	TEM sa 30 ! sets temperature of all surfaces to
	30°C
DEL TEM sij sa	Deletes temperature data for surfaces $sij$ or all surfaces (sa). The construction data are retained from the previous temperature state. For example, deleting temperature data on a lens at a higher tem- perature (say at 80°C), retains all construction data at the expanded temperature level. To restore the lens condition at room temperature (20°C), first ap- ply the command TEM sa 20 and then delete tem- perature data (DEL TEM sa).
EXC sij sa expansion_coef,or	
CTE sij sa expansion_coef	Linear expansion coefficient for mount, glasses or
	surface(s). The assumed exponent is $10^{-6}$ .
EXM sij sa expansion_coef	
	Linear expansion coefficient for first surface mir-
	ror substrate. The assumed exponent is $10^{-6}$ . Val-
	ues apply to the substrate for the designated sur-
	face(s) sij or all surfaces sa.
EXR sk sij ref_expansion_coef	Linear expansion coefficients for globally refer-
	enced distances. See also a detailed explanation
	below (section 21.1.2).
	Enter absolute $dn/dT$ values explicitly if the coef-
	ficients are unavailable in the glass catalogues. The
	assumed exponent is $10^{-6}$ The second form expects
	data in the order the system wavelengths are speci-
	fied. Thus, for 3 wavelengths defined, 3 dndt-values
	must be entered. The dndt-values must correspond
DNDT si jui dndt	to the system wavelengths. If there are more wave-
DNDT si $i$ dndt (w1)	lengths defined than dndt-values entered in the sec-
dndt (wn)	ond command form, $dn/dT = 0$ is assumed for the
	remaining wavelengths.
	Example 1: dndt s3 w15 -1.5
	Example 2: dndt s3 1.5 2.5 3.5
	See also querying DNDT as a LDI item (sect. 27,
	page 477. Further information on absolute and rela-
	tive dndT is given in sect. 13.2, page 223.
	continued on next page

continued from previous page	
DNDTC sij clc6	Enter $dn/dT$ coefficients for the surface(s) sij. The coefficients are $D_0, D_1, D_1, E_0, E_1$ in equation 13.17. Use of this command is recommended only where dn/dT data are not available in the catalogue glass model. Note, that in this command the coefficients are assigned to a specific surface and not to a catalogue glass, which is the normal case.

Changing the temperature causes all glass elements to expand or contract according to the expansion coefficient (EXC). Radii of curvature, axial thicknesses, aperture radii and aspheric coefficients change according to

$$L(T + \Delta T) = (1 + \alpha \cdot \Delta T) \cdot L_0 \tag{21.1}$$

where L is a length at the changed temperature, T is the base temperature,  $\Delta T$  is the change in temperature and  $\alpha$  is the linear expansion coefficient.

All air spaces are changed by computing the change in the corresponding *axial* thicknesses and adding the thickness change to the axial separation. In the case of strongly bent surfaces the length of spacers may significantly differ from the axial air space. In this case the correct spacer expansion must me modeled by auxiliary surfaces with appropriate CTE assignments.

For surfaces, which are globally referenced to a preceding surface, the reference thickness (THR) is changed according to the linear expansion coefficient EXR of the reference surface (see also section 21.1.2).

The expansion coefficient of the mount materials must always be explicitly entered using the EXC command.

The linear expansion coefficient of front surface mirrors must be explicitly entered by the EXM command.

Refractive indices change with the corresponding dn/dT-coefficient of the glasses. The dn/dT-coefficient is unique for each glass/material and is taken from the glass catalogues, if available. If not available, it is set to zero or it may be explicitly entered using the DNDT command.

## **21.1.1** Temperature Effects on "zoomed" Parameters (Multiconfiguration)

The thermal change of parameter defined in a Zoom/Multiconfiguration environment is also automatically adjusted with temperature, however, only a limited range of parameter is supported:

THI, THR

These two parameter allow the modelling of axial movements of components as is typical in classical variable focus lens systems.

## 21.1.2 Expansion Coefficients on Global References

In order to fulfil certain requirements on thermal behaviour of an optical system, for example athermalization, it is sometimes required to apply special mounting techniques where single lenses or groups of lenses are mounted in separated housings. Quite often, housing materials with abnormal thermal expansion coefficients are used to maintain focus without any powered drive mechanism (passive athermalization). When temperature changes, lenses (or lens groups) may move relative to another surface, typically a surface other than the immediately preceding one. The effect is that the change of the air space between two lenses is not dictated by the thermal expansion of the housing material, but follows a more complex relation.



Figure 21.1: Modelling thermal expansion with globally referenced surfaces.

Fig. 21.1 indicates a simple optical system, where the last lens (surfaces 7-8) is mounted in a separate housing being attached to a flange on the main housing close to surface 4. If the main housing and the sub-housing for lens 4 are made of different materials, the air space between the third and fourth lens will change according to the expansion difference of the two materials involved.

In order to adequately model this optical-mechanical configuration, surface 7 is globally referenced to surface 4. See also section 8.22 (page 118) for a general description of global references.

Instead of specifying the expansion coefficient of the air space between surfaces 6 and 7, we directly specify the expansion coefficient for the reference length surface 7 to surface 4. This is EXR, which always refers to a surface *before* the current surface. In other words, EXR is the linear expansion coefficient of a reference thickness (THR).

## 21.2 Pressure

A pressure profile may be assigned to a range of surfaces or to the entire lens system. Inhomogeneous pressure profiles in axial direction may be accomplished by assigning different pressures to different surface ranges.

PRE sij sa pressure	Pressure in mm Hg at surface(s) sij or all surfaces
	(sa). Example: PRE sa 760, sets the pressure to 760
	mmHg (normal pressure).
DEL PRE sij sa	Deletes pressure data for surfaces sij or all surfaces
	(sa).

## Tolerancing

22

The goal of any tolerancing scheme is to determine the dimensional ranges of optical components that meets performance requirements. Tolerances are variations in design data related to fabrication considerations. Careful tolerancing is important for the designer to ensure that the performance will be maintained in the finished units. The various tolerances may be used in any combination to evaluate the impact of fabrication errors. The tolerance perturbations for system prescription data are always taken from the currently assigned values. Tolerances are automatically saved with the lens file.

The two most common effects in tolerancing an optical system are underspecification, that is incompletely describing of what is required, and overspecification, wherein much more severe tolerances are established than required. Thus, defining tolerances is a complicated process between the limits imposed by

- a) the performance requirements of the optical system, and
- b) the expenditure of money and time which is justified by the application.

As a guideline, tolerances should be established as large as the requirement for satisfactory performance of the optical system will permit. The tolerancing calculations available in OpTaliX are divided into three separate categories:

- Sensitivity analysis
- Inverse tolerancing
- Monte Carlo analysis

All of these categories require the definition of *tolerance items* (section 22.1, page 407) and *tolerance criteria* (section 22.2, page 414, which are described in the following two sections.

## **22.1** Surface Tolerance Items

Tolerance items assigned to surfaces can be edited by the command EDI TOL, which invokes a dialog box, or they may be directly specified in the command line as described below. A detailed definition of each tolerance item is given in the table below and in the following sections.

EDI TOL	Opens a dialog box for editing surface tolerances.
DEL TOL [sij]	Delete all types of existing tolerances on designated sur- faces sij. Example: del tol s13 ! Delete tolerances at surface 1 to 3. del tol sa ! Delete tolerances at ALL surfaces.
DLF sij tol_testplate_fit	Tolerance on test-plate fit (in fringes at $\lambda = 546nm$ ) over the clear aperture. See also section 22.1.3 for more information. In ISO 10110 notation, DLF corre- sponds directly to the A-value, e.g. 3/ A (B, C) is synonymous to 3/ DLF (B, C). Note that sensitivity on test-plate fit may also be included in optimization us- ing the TSF function (see page 367). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.
IRR sij total_irregularity	Tolerance on cylindrical irregularity, in fringes at $\lambda = 546nm$ . The irregularity of a spherical surface is a measure of its departure from sphericity. See sect. 22.1.4 for more details. Note that sensitivity on surface irregularity may also be included in optimization using the TSI function (see page 367). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.
SYM sij symmetrical_irregularity	Tolerance on symmetrical aspherical irregularity, in fringes at $\lambda = 546nm$ . In ISO 10110 notation, SYM corresponds directly to the C-value, e.g. 3/ A (B, C) is synonymous to 3/ A (B, SYM).
DLT sij tol_thickness	Tolerance on axial thickness, in mm. Shows the effect of a change in the axial thickness between surfaces. Thick- ness tolerances applied to a surface will also move sub- sequent surfaces, except the subsequent surface(s) is/are globally referenced to any other preceding surface. See also sections 22.1.6 and 22.1.7 for more information. Note that sensitivity on surface irregularity may also be included in optimization using the TST function (see page 367). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.
DTR sij tol_ref_thickness	Tolerance on (global) reference thickness (see THR), in mm. Shows the effect of a change in the reference thick- ness. This option is only applicable for surfaces, which are globally referenced to a preceding surface. See also sections 22.1.6 and 22.1.7 for more information.
	continued on next page

DLN sij tol_index	Tolerance on index of refraction, at the reference wave- length. The tolerance value tol_index is specified as absolute difference to the nominal index. Example: dln s3 0.001 ! increases index of refraction by 0.001 Note that sensitivity on surface irregularity may also be included in optimization using the TSN function (see page 367). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.
DLV sij tol_V_number	Tolerance on dispersion. The tolerance value is speci- fied as a fraction of the nominal Abbe number $\nu_d$ . Example: dlv s3 0.008 ! changes the Abbe number by 0.8% Note that sensitivity on dispersion may also be included in optimization using the TSV function (see page 367). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.
DLR sij tol_radius	Tolerance on <i>absolute</i> radius, in mm.
HOM sij tol_homogeneity	Tolerance on index homogeneity, in $10^{-6}units$ . See also section 22.1.9, page 413 for details. Note that sensi- tivity on index homogeneity may also be included in op- timization using the TSH function (see page 368). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.
AXG sij tol_axial_grin	Tolerance on axial linear index gradient
RAG sij tol_radial_grin	Tolerance on radial quadratic index gradient
DLX sij tol_x_decenter	Tolerance on lateral displacement in X-direction, in mm. Note that sensitivity on X-displacement may also be in- cluded in optimization using the TSX function (see page 367). This option allows minimization of tolerance sen- sitivity on this parameter, whenever possible.
DLY sij tol_y_decenter	Tolerance on lateral displacement in Y-direction, in mm. Note that sensitivity on Y-displacement may also be in- cluded in optimization using the TSY function (see page 368). This option allows minimization of tolerance sen- sitivity on this parameter, whenever possible.
DLZ sij tol_z_decenter	Tolerance on longitudinal displacement in Z-direction, in mm. Note that DLZ is equivalent to a thickness toler- ance. Also note that sensitivity on Z-displacement may be included in optimization using the TSZ function (see page 368). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.

continued from previous page	
DLA sij tol_a_tilt	Tolerance on tilt about X-axis ( $\alpha$ -tilt), in arcmin. Note that sensitivity on tilt about X-axis may also be included in optimization using the TSA function (see page 368). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.
DLB sij tol_b_tilt	Tolerance on tilt about Y-axis ( $\beta$ -tilt), in arcmin. Note that sensitivity on tilt about Y-axis may also be included in optimization using the TSB function (see page 368). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.
DLG sij tol_c_tilt	Tolerance on tilt about Z-axis ( $\gamma$ -tilt), in arcmin. Note that sensitivity on tilt about Z-axis may also be included in optimization using the TSG function (see page 368). This option allows minimization of tolerance sensitivity on this parameter, whenever possible.

## 22.1.1 Tolerance Editor

Editing of surface tolerance items, tolerance criteria and compensators is accomplished from the menu Edit -> Tolerances or by clicking on the TOL button in the toolbar. A dialog box as shown in Fig. 22.1 is invoked.

📢 Toler	ances											X
	DLF	IRR	(	DLT		DTR	DLN		DLV		<u> </u>	Tolerance Functions
OBJ	0.00000	0.00000		).00000		0.00000	0.00000		0.00000			Limits
1	2.00000	0.40000	<b>~</b>	1.04000	<b>~</b>	0.00000	0.00050	~	0.00160	<b>∠</b>		MTPATT 1 Illean MTP (5+1)/2 - 5.0000
2	2.00000 🔽	0.40000		0.04000	~	0.00000	0.00000		0.00000			SPD f3 ! rms spot diameter _ 0.15000E-02
3	2.00000 🔽	0.40000	<b>v</b> (	).04000	<b>N</b>	0.00000	0.00050	~	0.00160	V		EFL ! equiv. focal length 💌 0.0
4	2.00000 🔽	0.40000	<b>v</b> (	).04000	ন	0.00000	0.00050	~	0.00160	4		CY si f1 w1 ! direction cosine Y 💌 0.0
5	2.00000 🔽	0.40000	V (	).04000	7	0.00000	0.00000		0.00000			
STO	0.00000	0.00000		).00000	Γ	0.00000	0.00000	-	0.00000			
7	2.00000 🔽	0.40000	<b>v</b> (	).04000	7	0.00000	0.00050	-	0.00160	1		
8	2.00000 🔽	0.40000	<b>v</b> 0	).04000	-	0.00000	0.00050	-	0.00160	1		Compensators
9	2.00000 🔽	0.40000	<b>v</b> (	).04000	2	0.00000	0.00000	-	0.00000			-
10	2.00000 🔽	0.40000	<b>v</b> (	0.04000	7	0.00000	0.00050	-	0.00160	1		() none
11	2.00000 🔽	0.40000	V (	).04000	7	0.00000	0.00000		0.00000			<ul> <li>back focus</li> </ul>
IMG	0.00000	0.00000		).00000	Γ	0.00000	0.00000	-	0.00000			C use settings defined in optimization
											_	
										ь ľ	~	🔽 Calculato pluo (minuo constituitu
										<u> </u>		<ul> <li>Calculate plus/minus sensitivity</li> </ul>
	elect default tole	erances										
0	🗅 None											
(	🗋 Low	Set										
(	🖲 High					C	ilear Tol.		Help			Cancel OK
(	) ISO 10110 d	efault										

Figure 22.1: Spreadsheet for editing surface tolerance items and tolerance criteria.

Surface tolerances are entered in rows (surfaces) and columns (tolerance type). Each tolerance must be made active in the check box right to each tolerance field. If the field is unchecked, it is not used in subsequent tolerance analyses.

Default tolerances in various grades may be assigned to surfaces (see section 22.1.2).

Up to eight performance criteria may be arbitrarily selected from the pull down menus. The example in Fig. 22.1 shows four performance criteria, which will be evaluated depending on surface or component tolerances:

MTFA f1	! mean MTF at field 1
SPD f1	! rms spot diameter at field 1
EFL	! equivalent focal length
CY si fl wl	! direction cosine Y at the image plane, field number 1 and wavelength
	number 1. This function gives a good measure of boresight stability.

The default setting for compensators is none.

#### 22.1.2 Default Tolerances

Default tolerances may be assigned to certain construction items. These tolerance values are taken from the ISO 10110-5 standard. Two other grades on tolerances are provided, "low" and "high", which are intended for "low"-performance and "high"-performance systems respectively.

It is important to note, however, that these default tolerances may not be appropriate for your particular optical performance requirements. Therefore, the defaults should be considered as convenient starting points for examining the relative sensitivities of the various lens parameters. It is up to the user to deviate from the defaults and change the tolerances correspondingly.

#### 22.1.3 Tolerance on Test-Plate Fit (DLF)

Shows the effect of a change in the radius of curvature of a surface. The perturbation is specified in terms of interference fringes<sup>1</sup> relative to test plate or interferometer fit at the *reference wavelength* used in the optical system. As default, ISO 10110-5 specifies  $0.54607\mu m$  (e-line). If the reference wavelength differs from  $0.54607\mu m$ , the tolerance specification may be converted to another wavelength by

$$DLF_{\lambda 2} = DLF_{\lambda 1} \cdot \frac{\lambda_1}{\lambda_2} \tag{22.1}$$

where  $DLF_{\lambda 1}$  and  $DLF_{\lambda 2}$  are the numbers of fringe spacings at  $\lambda_1$  and  $\lambda_2$ , respectively.

The number of fringe spacings corresponding to a dimensional radius tolerance, provided the radius change is small, is given by

$$DLF = \frac{2\Delta R}{\lambda} \left[ 1 - \sqrt{1 - \left(\frac{D}{2R}\right)^2} \right]$$
(22.2)

If the ratio D/R is small, Eq. 22.2 may be approximated by

$$DLF = \left[\frac{D}{2R}\right]^2 \frac{\Delta R}{\lambda} \tag{22.3}$$

Note that in ISO 10110-5 notation, DLF corresponds directly to the A-value, e.g. 3/A (B, C) is synonymous to 3/DLF (B, C). More generally, 3/A (B, C) is equivalent in OpTaliX to 3/DLF (IRR, SYM).

<sup>&</sup>lt;sup>1</sup>Due to the double pass of test plate or interferometer tests, fringes give twice the surface error measured in waves.

## 22.1.4 Tolerance on Irregular Surface Deviation (IRR)

Tolerance on cylindrical irregularity, in fringes at  $\lambda = 546nm$ . The irregularity of a spherical surface is a measure of its departure from sphericity, that is a difference in the radii of curvature between the X/Z and Y/Z meridians. The irregularity is applied by increasing the value of the X/Z radius by  $\Delta R/2$  and by decreasing the value of the Y/Z radius by  $\Delta R/2$ .

In ISO 10110 notation, IRR corresponds directly to the B-value, e.g. 3/A (B, C) is synonymous to 3/A (IRR, C).

In statistical tolerance simulations (TOL STAT command, see also sect. 22.7), the orientation (azimuth) of the cylindrical deformation is assumed always along the local Y-coordinate axis.

## 22.1.5 Tolerance on Symmetrical Aspherical Surface Deviation (SYM)

The SYM tolerance specifies the rotationally symmetrical (aspherical) surface irregularity according to the ISO 10110-5 norm. As such, the SYM tolerance is directly comparable to the C-value in ISO 10110-5. More generally, 3/A (B, C) is equivalent in OpTaliX to 3/DLF (IRR, SYM).

In OpTaliX, SYM is modeled by a Zernike deformation using coefficient 9 (spherical and focus,  $3^{rd}$  order) to generate a surface deformation of SYM fringes. Example: SYM 1.0 (fringes) corresponds to a PV surface deformation of 0.000273 mm at the reference wavelength 546nm. A representation of this error form is given in Fig. 22.2.



Figure 22.2: Symmetrical (aspherical) surface deformation representing the ISO 10110 C-value.

## 22.1.6 Tolerance on axial Thickness (DLT)

Axial thickness tolerances (DLT) change both, thicknesses of lens elements and of air spaces between lenses. The way DLT-tolerances affect the optical system depends on how subsequent surfaces are referenced. Fig. 22.3 shows the effects of DLT for two cases:

- a) All surfaces are sequentially referenced, that is the position of a surface is defined with respect to its immediately preceding surface. A thickness tolerance of the first surface (DLT s1) will move the absolute position of all subsequent surfaces.
- b) Surface 3 is globally referenced to surface 1. A thickness tolerance of the first surface does not change the absolute position of subsequent surfaces (here surfaces 3 and 4) and surface 2 now moves into the air space between the first and second lens.



Thus, in order to apply tolerance changes to the absolute position of surface 3, a DTR-tolerance must be assigned to this surface.

Figure 22.3: Axial thickness tolerance for different types of surface referencing.

#### 22.1.7 Tolerance on global Thickness (DTR)

A DTR-tolerance changes the axial position of a surface, which is referenced to a preceding surface. This must not be confused with a DLT-tolerance at the same surface. As for the nominal value THR, which defines the separation *before* the surface vertex to the referenced surface, the DTR-tolerance changes the nominal THR value.

Since a surface may be globally referenced to another surface, which itself is globally referenced (i.e. a chain of global references), complex housings and interdependencies can be simulated. Referring to Fig. 22.3b, we see that surfaces 1 and 3 are directly attached to the housing. Since tolerances on mechanical distances are generally different from tolerances on lens thicknesses, also DLT and DTR tolerances will be different.

#### 22.1.8 Tolerance on Surface Tilt (DLA, DLB, DLG)

Tolerances on surface tilts are expressed by DLA, DLB, DLG, representing the tilt around the x-axis, y-axis and z-axis, respectively. The tilt tolerances are defined in minutes of arc (arcmin). This unit has been chosen to directly relate to typical drawing specifications about tilt and lens wedge.

## 22.1.9 Tolerance on Homogeneity (HOM)

Homogeneity of refractive index (HOM) is modelled in OpTaliX by a radially symmetric gradient, which cannot be completely cancelled by a focus compensator. The radial GRIN model used is

$$n = n_0 + c_t r^2 (22.4)$$

where  $n_0$  is the base (vertex) index of the glass, r is the radial distance from the optical axis and  $c_t$  is calculated from the specified index tolerance  $\Delta n = n - n_0$ . Note that  $\Delta n$  must be specified in  $10^{-6}$  units.

## 22.2 Tolerance/Performance Criteria

Once reasonable tolerances are entered, *tolerance criteria* are established to allow a sensitivity tolerance analysis based on any quality measure available in OpTaliX. Tolerance criteria are measures of system performance, whose sensitivities to changes in the construction parameters we wish to study. Thus, a tolerance function may be any arbitrary performance measure such as rms-spot diameter, MTF, Strehl ratio or boresight, to name a few. Anything that can be computed as an performance measure and that can be addressed in the optimization can also be used as a criterium in tolerance analysis. An overview of available performance functions is found in section 19.7, page 363. This approach provides the capability to "tolerance on anything".

TOLC fcn_no fcn_string	Tolerance criterium, i.e. the performance measure to be used in sensitivity analysis. Up to 5 tolerance criteria can be simultane- ously defined for sensitivity analysis. fcn_no is the number of the function (criterium), which must be between 1 and 5. Toler- ance criteria may also be edited in a dialog box, which is invoked by EDI TOL. Since tolerance criteria usually contain blank characters, fcn_string must be enclosed in apostrophes if entered in the command line. Examples: tolc 2 'spd f3' ! Defines rms spot diameter at field 3 as tolerance criterium. It is stored as $2^{nd}$ function. tolc 3 'mtfa f3' ! Defines average (mean) MTF at field 3 as tolerance criterium. Note, that MTF is always given in %, ranging between 0 and 100.
TOCL fcn_no limit	Limit on tolerance criterium, to be used in inverse sensitivity anal- ysis. fcn_no is the number of the function (criterion), which must be between 1 and 5. Example: tocl 3 5 ! In the second example of the TOLC command (tof 3 'mtfa f3') a degradation limit of 5% is defined for mean MTF at field 3. Note that MTF is always specified in %.

## 22.3 Tolerance Compensators

Compensators are variable construction parameters that are changed after a tolerance has been applied. The most common compensator is the back focus to keeping the image plane always at best focus, but also any other parameter may be used to adjust for arbitrary performance measures.

The introduction of compensators prior to calculating tolerances is an important means for reducing tolerance sensitivity of an optical system. There are two basic compensation methods:

a) Adjusting the back focus only,

b) defining a complete optimization set, which may have multiple compensating variables.

TOCM NO BF OPT TOlerance BF uses OPT use	Tolerance compensator method.
	NO disables compensator,
	BF uses back focal length as compensator (see section 22.3.1),
	OPT uses settings in optimization as compensator (see section 22.3.2).

Tolerance compensators can be specified by the command

#### 22.3.1 Back Focus Compensator

Adjustment of the back focus is performed by the autofocus module. By default, minimum rmsspot size at all fields and wavelengths is used for finding the optimal focus. If focus adjustment for selectable fields, wavelengths or other performance criteria is desired, optimization shall be used as compensating module (see below).

## 22.3.2 Compensation using Optimization

Arbitrary construction parameter and target (performance) criteria may be selected when tolerance compensation is performed via the optimization module. This requires proper setting of variables and performance criteria. The optimization settings may be identical to the settings used for optimization of the system. Compensators are designated by optimization variables (i.e. thicknesses, radii of curvature, etc). However, it is preferable to setup special optimization settings, since generally only a few parameters (for example air spaces) will be used for tolerance compensation.

Before using the tolerancing routines, make sure that the current optimization variables correspond to those system parameters that you wish to use as compensators. See section 19, page 349 for defining optimization variables and performance functions (criteria).

Using optimization is much more powerful than simply adjusting the back focus, as any construction parameter, which can be edited, can be used as a compensator. There is also no limit in the number of compensator variables. Typical compensator variables used in tolerancing are air spaces and lens/group tilts or decentrations.

The functions (performance criteria) defined and used in the optimization module are completely independent from the tolerance criteria (section 22.2). Thus, it is possible to compensate (optimize) on wavefront and analyse tolerance sensitivity on MTF.

## 22.4 Sensitivity Analysis

This analysis provides information about the direct sensitivity of an optical system to fabrication and mounting errors. Each parameter is changed by its tolerance, and the changes in the requested performance measures are computed.

TOL SEN	Performs a sensitivity analysis based on surface tolerance items and toler-
	ance criteria, both defined under EDI TOL

The variation of most performance measures is, in general, approximately quadratic with respect to changes of lens (construction) parameters. To model this variation, sensitivity is calculated for plus and minus tolerances and a quadratic function F as given in Eq. 22.5 is then calculated.

 $F = A \cdot T^2 + B \cdot T + C \tag{22.5}$ 

For each individual pair of tolerance and performance criterion a quadratic equation is calculated. For example, 5 types of tolerances at 10 surfaces and three tolerance/performance criteria will already create  $5 \times 10 \times 3 = 150$  quadratic functions.

Once surface tolerance items (section 22.1) and tolerance criteria (section 22.2) are established, a sensitivity analysis can be run. As an example, we use the Cooke triplet from the examples library \optix\examples\misc\cooke.otx. For the sake of simplicity, we only define tolerances on test-plate-fit, irregularity, axial thickness and x-decenter at the first three surfaces. The axial shift of the focal surface (back focus) is used as compensator. It is worthwhile to remember that back focus adjustment uses the autofocus module, which - by default - optimizes for minimum spot size over the entire field. This may or may not be appropriate for a specific application. Other compensators may be defined in the optimization settings (see sections 22.3.2 and 19). We will also define three tolerance criteria, the on-axis MTF and the tangential and sagittal MTF separately at field number 2, which is at 70% of the maximum field. These are the system performance measures, whose sensitivities to changes in the construction parameters we wish to study.

TOLERANCE DATA : 3.0000 DLF s1 IRR sl 2.0000 DLT s1 0.10000 DLX s1 0.50000E-01 DLF s2 3,0000 s2 2.0000 IRR 0.10000 DLT s2 DLX s2 0.50000E-01 DLF s3 3.0000 IRR s3 2.0000 0.10000 DLT s3 DLX s3 0.50000E-01 Compensator: back focus. Tolerance Criteria: MTFA f1 ! mean MTF (S+T)/2 MTFT f2 ! tangential MTF MTFS f2 ! sagittal MTF

The sensitivity analysis is started with the command "SEN" or by selecting *Manufacturing* –> *Tolerances* –> *Sensitivity analysis* from the main menu.

```
TOLERANCE SENSITIVITY ANALYSIS
Compensator: back focus (BFL)
                               MTFT f2
                     MTFA fl
                                          MTFS f2 BFL-Change
Nominal value(s)
                     91.62532
                                          35,41631
Sur Tol. (fringes)
 1 DLF 3.0000 (+)
                    0.19083
                               -1.31205
                                        1.72375
                                                    0.00244
                                                    0.01047
                              -0.43768
                     0.38478
                                           1.98080
              (-)
 2 DLF 3.0000 (+)
                      0.37379
                                           1.40129
                               0.42367
                                                     0.01046
                     0.13386 -1.94613
                                           1.81060
                                                    0.00080
              (-)
 3 DLF 3.0000 (+)
                    -0.05128
                               -1.11433 0.85838 -0.01033
                    0.51189 -0.77738
                                          2.93915
                                                    0.02351
               (-)
           RSS
                    0.77896
                               2.77957
                                           4.63812
Sur Tol. (fringes)
                                                     0.02389
                     -0.14500
                               -3.56583
 1 IRR 2.0000 (+)
                                        -3.22650
               (-)
                     -0.12578
                                1.52675
                                           7.49339
                                                     -0.00928
 2 IRR 2.0000 (+)
                     -0.14084
                                1.75238
                                           7.72477
                                                     -0.00927
                    -0.19613
                               -3.71870 -3.59981
                                                     0.02318
              (-)
 3 IRR 2.0000 (+)
                     -1.64383
                               -6.54326
                                          -7.60950
                                                     0.04369
                     -1.76839
                                        12.38967
              (-)
                               4.15559
                                                     -0.02792
```

		RSS		2.43403	9.59317	18.72432	
Sur	Tol.	(mm)					
1	DLT	0.1000	(+)	0.33377	-1.69334	2.79460	0.01194
			(-)	0.24226	-0.07476	0.85278	0.00087
2	DLT	0.1000	(+)	0.48737	4.42504	2.10420	0.03149
			(-)	-0.58395	-5.42251	0.79647	-0.02039
3	DLT	0.1000	(+)	-0.56635	-7.47778	2.78950	-0.01111
			( – )	0.52615	6.20604	-0.76605	0.01977
		RSS		1.16026	12.09503	4.68692	
Sur	Tol.	(mm)					
1	DLX	0.0500	(+)	0.03605	-1.48804	1.98951	0.00730
			(-)	0.03597	-1.48800	1.98886	0.00729
2	DLX	0.0500	(+)	0.29881	-0.98564	1.93998	0.00706
			( – )	0.29878	-0.98563	1.93977	0.00706
3	DLX	0.0500	(+)	-3.09337	-2.01578	-1.17260	0.01254
			( – )	-3.09320	-2.01357	-1.17472	0.01255
		RSS		4.39522	3.80646	4.26555	
	То	tal RSS		5.21493	16.14106	20.30455	

At the top of the sensitivity table (sometimes called change table) are the nominal values of the tolerance criteria, that is the performances of the undisturbed system. The output is grouped in the different types of tolerances (e.g. test-plate-fit, irregularity, etc) and within each group tabulated according surface numbers. Each column lists the *changes* in MTF for each tolerance item.

The changes in the back focus compensation are listed in the rightmost column under the label "BFL-Change". If more than one tolerance criterion is defined, the maximum value of back focus compensation is printed. The RSS values given for each column and each tolerance group is a "statistical sum" of the performance perturbations  $\Delta F$  and is defined as

$$RSS = \sqrt{\Delta F^2} \tag{22.6}$$

Tolerance sensitivities are usually given for plus and minus tolerances respectively. This is indicated by (+) and (-) in the sensitivity table.

## 22.5 Tolerance Sensitivity in Optimization

Typically, an optical designer needs to find the optimal compromise between optical performance, costs, volume constraints and manufacturing aspects. In particular, the latter requirement asks for an optical system that is insensitive to manufacturing tolerances to a maximum extent.

That is, optimizing for maximum (optical) performance alone will most likely not yield a design that fulfills all requirements mentioned above. Furthermore, considering the sequence of a typical design process, we have concept design, optimization, tolerancing and then, if needed, several re-iterations to achieving a design that can be economically manufactured.

This is a tedious process. OpTaliX helps you in that it allows integration of tolerancing issues already during the optimization process. This means that you can specify certain surfaces (or all surfaces) whose sensitivity to alignment errors or manufacturing errors in general are to be minimized. Thus, in other words, OpTaliX can simultaneously optimizes for both optimum image performance and minimum tolerance sensitivity.

See the commands TSF, TST, TSI, TSN, TSV, TSX, TSY, TSZ, TSA, TSB, TSG for defining tolerance sensitivity functions in optimization (sect. 19.11 and pages 367 to 368).

Tolerance sensitivity is calculated on the basis of wavefront aberration (WAV) for a given tolerance item. A basic introduction to the method used in OpTaliX is given by Grey [16], and practical examples are given by Isshiki et.al, [23].

## 22.6 Inverse Tolerancing

Inverse tolerance analysis starts from a predefined change in system performance and determines the tolerance limit for each construction parameter. This analysis is based on the functional relationship between tolerances and performance measures, which is obtained during sensitivity analysis from the quadratic functions in Eq. 22.5. Then, using this data, the allowed tolerances for specified changes in performance (the tolerance criteria) are computed.

TOL INV	Performs an inverse tolerance based on tolerance criteria (TOLC) and limits
	on tolerance criteria (TOCL), both defined under EDI TOL

## 22.7 Monte Carlo Analysis

The Monte Carlo tolerancing is a statistical approach to simulate production yields on the basis of predetermined surface/component tolerances. It allows prediction of freely definable performance metrics on the basis of statistical (random) perturbations of construction parameters within limits defined by the individual surface/element tolerances.

A successful statistical tolerance (yield) analysis is performed in several steps:

- Define the surface/component tolerances, e.g. in the tolerance editor (22.1.1), tab "Tolerances".
- Define the performance parameters you want to analyze, e.g. in the tolerance editor (22.2), tab "Tolerance Functions".
- Define the statistical distributions of tolerances and the statistical population (number of individual objectives), e.g. in the tolerance editor (22.7.1), tab "Statistics".
- Run the statistical analysis, e. g. by the command TOL STAT or from the tolerance dialog, tab "Analyses".

A central dialog allows defining and editing of all tolerance parameters and function. It is invoked by the command EDI TOL, or from the main menu "Edit" -¿ "Tolerance Editor".

#### 22.7.1 Statistical Parameters and Distributions

The parameter variation within a given tolerance can be differently distributed. Currently, three distribution forms are possible:

- Even distribution
- Gaussian distribution
- Beta distribution



Figure 22.4: Even distribution with pseudo-random numbers. Left: linear plot, right: cumulative plot.

#### 22.7.1.1 Even Distribution

This distribution form assumes that all parameter perturbations are evenly distributed within a given maximum tolerance. A graphical illustration is given in Fig. 22.4 below.

#### 22.7.1.2 Gaussian Distribution

The Gaussian distribution is the most common form in statistical tolerancing. The statistical perturbations are based on normally (Gaussian) distributed pseudo-random numbers with zero mean. In OpTaliX tolerancing, the Gaussian distribution accepts one parameter  $\sigma$  which denotes the standard deviation. For  $1\sigma$  about 68% of all perturbations lie within the tolerance band defined,  $2\sigma$  will include 95.4%, and  $3\sigma$  include 99.7% of all tolerance perturbations.



Figure 22.5: Gaussian distribution with  $2\sigma$  variance on a  $\pm 0.1mm$  tolerance. Left: linear plot, right: cumulative plot.

## 22.7.1.3 Beta Distribution

The Beta distribution is a special continuous probability distribution that allows simulation of special non-symmetrical distributions. It is currently implemented with fixed parameters ( $\alpha = 2, \beta = 5$ ) that result in the distribution form given in Fig. 22.6.

This distribution is well suited to modeling fabrication specific effects. For example, polishing/grinding of lenses is typically stopped when the thickness of a specific lens is within a defined

tolerance. Because this process always starts from a thicker blank and removal of material reduces the axial thickness, there is a tendency that axial thicknesses of lenses towards the upper tolerance interval, hence, the non-symmetrical thickness distribution.



Figure 22.6: Beta distribution. Left: linear plot, right: cumulative plot.

## 23

## **Manufacturing Support**

## 23.1 Footprint Analysis

The footprint option plots the boundaries of the light beams going through the optical system on a specified surface. This is done by calculating the intersection of the beam with the surfaces of interest. In case of curved surfaces, the beam intersections are plotted parallel to the local Z-axis onto the vertex tangent plane. All wavelength, activated fields and zoom positions are represented and the resulting plot is a composite of the used area of the surface. Vignetting is always taken into account. Note that rays are only vignetted if a fixed aperture (see FHY command, page 171) has been assigned to the designated surfaces. Internal obscurations are not taken into account in footprint analysis. They are, however, considered in the ray intersection analysis (page 14.1.8), which is equivalent to footprint analysis, where a ray grid is traced to the designated surface.

	Plot the footprint or	n surface sk for fields fij. For			
	'zoomed' (multi-configuration) systems, the currently selected				
	zoom position is use	d (see POS command). The parameter			
	plot_extent is opt	ional and defines the maximum displayed			
	area. Absence of plo	ot_extent or a zero value invokes au-			
	tomatic determination	of the plot area on sk, respectively uses			
	the previously entered	l value of plot_extent. The optional			
	parameter NUM outpu	its additional data, such as enclosed area,			
	center of gravity and	maximum extensions of the beam foot-			
FOO [sk   fij	prints (see page 23.1).				
plot_extent NUM ? ]	Examples:				
	FOO	plots the footprint for all fields. Sur-			
		face 1 is the default.			
	FOO ?	invokes a dialog box to select sur-			
		face, field and plot extents.			
	FOO s4 f46	plot footprint on surface 4, fields 4			
		to 6.			
	FOO s4 25.0	footprint with manual definition of			
		plot_extent, all fields.			

Like many options in OpTaliX, for footprint analysis the chief rays must be traceable, even if it is obscured. Boundary calculations are performed by a search algorithm moving from the chief ray outward in radial direction until the stop aperture or a fixed aperture on any other surface in the system is found. The algorithm is not designed to handle obscuring sub-apertures like spiders, which divide the pupil into three (or four) parts.

See also the ray intersection option (page 14.1.8), which plots the used area on surfaces based on a full grid of rays traced to the selected surface for each field bundle and zoom position.

In the following example (Fig. 23.1), a fold mirror has been added behind a Double Gauss lens. The footprint on the fold mirror shown for nine field points indicates how large it must be to avoid additional vignetting of the beams within the field of interest.



Figure 23.1: Beam footprints on fold mirror behind a Double Gauss lens.

#### NUM Option in Footprints:

The NUM option in footprint analysis outputs additional data, such as enclosed area, center of gravity and maximum extensions of each beam footprint, separated for field and zoom position. Note that this analysis does NOT include aperture obscurations on the designated surface. See the sample output below:

FOOTP	RINT DATA	on Surface	1					
Pos.	Field	X-Center	Y-Center	Area (mm^2)	X-min	X-max	Y-min	Y-max
1	1	0.0000	0.0000	313.57982	-9.994	9.994	-9.994	9.994
1	2	0.0000	-4.1785	306.45888	-9.996	9.996	-13.943	5.578
1	3	0.0000	-9.3060	251.48431	-10.006	10.006	-16.999	-2.024
					-10.006	10.006	-16.999	9.994

## 23.2 Aspheric Deformation

The aspheric deformation option calculates the deviation of an aspherical (non-spherical) surface with respect to a perfect sphere. The radius of the perfect sphere is taken as a reference and can be selected according to different criteria.

Aspheric deformation is expressed as difference of the sag of the asphere to the sag of the perfect sphere (i.e. the reference sphere).

	Aspheric deformation in radial direction. Plots and prints the sag of the asphere compared to a reference sphere which may be contacting at one or two zones on the air side of the surface.sksurface number refrefreference describing the type of refer- ence radius, where ref can be one of:
ASD sk [ref] [ref_rad] [?]	VER : vertex radius CEN : center and rim zero RIM : only rim zero BFR : best-fit radius. ref_rad spherical reference radius
	Example:
	ASD s3 CEN : Plots aspheric deviation with
	reference radius calculated for zero deviation at
	center and rim of surface.
ASD2 [sk ?] [ref_rad]	Aspheric deformation shown over full surface area. The deformation is based on the reference radius ref_rad. If ref_rad is omitted or is 0, the vertex radius of the designated surface is used.

## 23.2.1 Aspherization in radial Direction

Enter "ASD ?" in the command line or select from the main menu *Manufacturing* - > *Aspheric Deformation* - > *in radial direction*. Four options are selectable in a dialog box to determine the reference radius

- 1. the vertex radius is taken as the reference radius
- 2. the reference sphere contacts center and rim of the surface
- 3. only the rim of the surface is contacted by the reference sphere,
- 4. a "best fit" approach is attempted (the reference sphere touches the aspheric surface at 0.7 of the aperture radius.

Each of the options has its distinct advantages. The following treatment shall be a concise guide in selecting the optimum reference radius (see figure 23.2).

#### Option 1:

Vertex Radius: This option is probably the first and simplest choice as it directly reflects the mathematical definition of the asphere. However, for fabrication purposes, it is not reasonable as the amount of material to be removed is extremely large. In addition, it may lead to infeasible solutions for steep (conic) aspheres, as already shown in the drawing above.

## **Option 2:**

Center + Rim Zero: The spherical reference radius is constructed such that the reference sphere has contact (touches) the asphere at two zones: The center (of revolution) and the rim (at the max. aperture). Thus, only in the intermediate zones, material must be removed.

#### **Option 3:**

Only Rim Zero: Here, the reference sphere touches th asphere at only one zone, the rim. Compared to option 2 (center and rim zero), much more material must be removed during grinding and polishing. The main advantage is, however, that the edge does not require further shaping during the subaperture grinding phase which generally avoids the "turned down edge" problem.

#### **Option 4:**

Best Fit: This option is equivalent to option 3 (only rim zero) but differs in that the zone at which the reference sphere touches the asphere is at 0.7 of the maximum aperture radius. Much less material must be removed (compared to option 3) but the danger of turned down edges during polishing exist.



Figure 23.2: Construction of reference radius to an aspheric surface.

In addition to the aspheric deviation plot, numerical values are also printed at 21 positions along the Y-height of a surface. A typical output lists the surface parameters (curvature, conic constant, aspheric coefficients) and subsequently the Z-coordinates at various radial heights in Y-direction.

[h] ASPHERIZATION DATA:

File : F15_33.0 Surface : 15	OTX	
Vertex Curvature	:	-0.17277313E-01
Vertex Radius	:	-57.87937061E+00
Conic Constant	:	0.0000000E+00
A	:	10.77564552E-06
В	:	23.69965431E-09
С	:	-53.48477648E-12
D	:	441.68107450E-15
E	:	0.0000000E+00
F	:	0.0000000E+00
G	:	0.0000000E+00
Н	:	0.0000000E+00

Aspherization is determined for zero deviation at center and rim. Radius = -91.49306

Radial heig	jht Z-Sphe	re Z-Asphere	e Difference	Slope		Surface Normal	
(1	nm) (n	m) (mm)	(mm)	(micron/mm)	CXN	CYN	CZN
0.000	0.0000	00 0.000000	0.000000	0.00	0.000000	0.000000	1.000000
0.700	-0.0026	78 -0.004231	-0.001553	-2.22	0.00000	0.012079	0.999927
1.400	-0.0107	12 -0.016893	-0.006181	-6.61	0.000000	0.024069	0.999710
2.100	-0.0241	03 -0.037897	-0.013794	-10.88	0.00000	0.035878	0.999356
2.800	-0.0428	55 -0.067093	-0.024238	-14.92	0.000000	0.047410	0.998876
3.500	-0.0669	69 -0.104261	-0.037291	-18.65	0.000000	0.058560	0.998284
4.200	-0.0964	52 -0.149108	-0.052657	-21.95	0.000000	0.069219	0.997601
4.900	-0.1313	06 -0.201261	-0.069955	-24.71	0.000000	0.079263	0.996854
5.600	-0.1715	40 -0.260255	-0.088715	-26.80	0.00000	0.088557	0.996071
6.300	-0.2171	59 -0.325522	-0.108363	-28.07	0.000000	0.096949	0.995289
7.000	-0.2681	73 -0.396376	-0.128204	-28.34	0.000000	0.104264	0.994550
7.700	-0.3245	89 -0.471991	-0.147401	-27.43	0.00000	0.110291	0.993899
8.400	-0.3864	19 -0.551366	-0.164947	-25.07	0.00000	0.114768	0.993392
9.100	-0.4536	73 -0.633286	-0.179614	-20.95	0.00000	0.117354	0.993090
9.800	-0.5263	63 -0.716246	-0.189883	-14.67	0.00000	0.117587	0.993063
10.500	-0.6045	02 -0.798349	-0.193847	-5.66	0.000000	0.114832	0.993385
11.200	-0.6881	04 -0.877160	-0.189056	6.84	0.00000	0.108190	0.994130
11.900	000 -0.7771	85 -0.949495	-0.172310	23.92	0.000000	0.096392	0.995343
12.600	-0.8717	60 -1.011118	-0.139358	47.07	0.00000	0.077646	0.996981
13.300	000 -0.9718	47 -1.056340	-0.084493	78.38	0.000000	0.049448	0.998777
14.000	000 -1.0774	64 -1.077464	0.00000	120.70	0.00000	0.008382	0.999965

The meaning of the columns is:

Z-Sphere	Z-coordinate of the base sphere, respectively the reference sphere if fit-
	ting to the deviation at the rim or to the best-fit sphere (options 2-4, see
	above) is requested.
Z-Asphere	Z-coordinate of the aspheric surface
Difference	The deviation of the aspheric surface from a sphere (either base sphere
	or best-fit sphere)
Slope	The derivative of the aspheric deformation with respect to the base or
	reference sphere, as shown in Fig. 23.3.
CXN, CYN,	Direction cosines of the surface normal.
CZN	



Figure 23.3: Slope of aspheric deformation based on the reference sphere.

#### 23.2.2 Aspherization as 2D Surface Deformation

Enter "ASD2 ?" in the command line or select from the main menu *Manufacturing* - > Aspheric*Deformation* - > as 2*D*-surface deviation which invokes a dialog as shown in Fig. 23.4.

👫 Aspheric Deviation
Surface 10 ★ Show as Wire grid ▼ Grid X: 32 ★ Y: 32 ★
Plot Scale 0.0000000 (0=automatic)
Reference radius -360.5000000 (0=automatic)
Show absolute surface shape
I Export deviation data to file
File: c:\temp\surface10.dat Browse
In global coordinates
Cancel OK

Figure 23.4: Dialog box for creating 2D surface deformation plots.

The program searches for the first aspheric surface in the optical system and displays the corresponding surface parameter in the dialog. The reference radius is always the vertex radius, however, it may be changed to any other arbitrary value.

2D aspheric deformation data may also be exported as X-Y-Z coordinates to a file in ASCII or Excel format. Note that this option is currently only available from the dialog.

## 23.3 Hologram Phase

This section displays the phase on diffractive surfaces, and indicates the required surface profile on a substrate according to the hologram coefficients.

HPH [?]	Plots phase on diffractive/holographic surfaces. Also plots the sag of the surface profile based on the corresponding hologram coefficients.
HPHN sj xabs yabs	Returns the phase (in waves) on a diffrac- tive/holographic surface sj. The parameter xabs, yabs are the local absolute coordinates (in mm) on this surface.
HZO [?]	Calculates the radial zones of radially symmetric diffractive (HOE) phase profiles based on $2\pi = 1\lambda$ intervals. Output is only generated on "H" and "G" surface types. Otherwise, an error message is displayed. See also sect. 23.3.2

### **23.3.1** Converting Symmetric Hologram Coefficients to other Programs

#### 23.3.1.1 To Code V

On hologram surfaces with symmetric phase functions, the OpTaliX hologram coefficients are converted to Code V by the following relation:

$$c_{CodeV} = \frac{c_{OpTaliX} \cdot \lambda_0}{1000}$$
(23.1)

Note that the factor in the denominator describes the conversion from micrometers (OpTaliX default) to nanometers (Code V default).

#### 23.3.1.2 To Zemax

The BINARY\_2 surface type in Zemax is a direct equivalent of symmetrical hologram surface in OpTaliX. The symmetrical hologram coefficients from the Zemax BINARY\_2 surface to OpTaliX are converted by:

$$c_{OpTaliX} = \frac{c_{binary2}}{2\pi \cdot R_N^i} \tag{23.2}$$

where  $R_N$  is the normalization radius in Zemax and *i* is the *i*<sup>th</sup> power of the coefficient. Note that the import may fail, because Zemax supports coefficients up to the  $i = 480^{th}$  power whereas OpTaliX is limited to coefficients of  $27^{th}$  power.

Other hologram (binary) surface types available in Zemax are not supported yet.

#### 23.3.2 Hologram Zone Calculation

This section describes calculation of zones on diffractive structures (in absolute and  $2\pi$  terms) with symmetrical phase profiles. The absolute phase is usually represented by a surface profile similar to Fresnel zones, where the steps are arranged at modulo  $(2\pi)$  phase intervals. Each interval corresponds to  $1\lambda$  phase difference at the reference (design) wavelength. A typical cross-sectional representation of the phase profile is given in Fig. 23.5.

The sagitta of the radial groove profile (i.e. modulo  $(2\pi)$  of the diffractive phase function), also commonly described as blaze depth d, is then calculated by [62],

$$d = \frac{\lambda_0}{n_0 - 1} \tag{23.3}$$

where  $\lambda_0$  is the reference wavelength, and  $n_0$  is the refractive index at the reference wavelength. The radial coordinates of rotationally symmetric diffraction zones are calculated by the HZO command. Phase  $2\pi$  steps are located at 1nm intervals which should be sufficiently accurate for all manufacturing aspects.

## 23.4 Edge Thickness

ET sij X_height Y_height	Edge thickness of surface(s) sij at surface co-
	ordinates X_height, Y_height. If X_height,
	Y_height are omitted, the clear aperture Y-height will
	be used. For tilted/decentered surfaces see the conven-
	tion in sect.23.4.1 below.



Figure 23.5: Modulo  $2\pi$  zones on diffractive surface with radially symmetric phase function

## 23.4.1 Calculating edge thickness at tilted/decentered surfaces

If any surface within of the specified range si..j is tilted or decentered, edge thickness (ET) is calculated with reference to the local coordinate system of the first surface in the range given, i.e. ET is measured along the local Z-axis of the first surface.



Figure 23.6: Edge thickness at tilted surfaces.

## 23.5 Test Plate Fitting

Performs automatic fitting of surface radii to a test plate list of a specific manufacturer. All test plate information is provided by the respective vendors.

TPL [sij   manuf]	Find the nearest radius of curvature from a manufacturers test
	sion manuf describes the manufacturer. The first three charac- ters are significant. See table 23.1 below for a complete list of
	available test plate lists. If manuf is absent, a dialog box will
	be opened.
	Example:
	tpl s47 ROD selects test plates from Rodenstock and re-
	places the actual radii of surfaces 4 to 7.
LIS TPL [manuf]	Reports test plate list of manuf. The first three characters of
	the manufacturer string are significant to identify the list. If
	manuf is omitted, a dialog box will be invoked for selection of
	the appropriate manufacturer.
	Examples:
	lis tpl mel
	lis tpl melles griot

## 23.6 Adding a Test Plate List

Test plate lists (TPL) are stored in readable unformatted ASCII files, ending in the extension TPL. New lists may be added easily if the specific TPL file structure is preserved. A detailed description of the test plate file structure is given in section 32.6.

The file "tplinfo.txt" in the ./testplat directory contains a summary of all available testplate files and a short description. New (user defined) testplate files must have an entry to this file. For each testplate list, two kinds of information must be entered (unformatted) in a single line, separated by at least one blank character:

The testplate filename (including extension) and a descriptive text to the testplate list, which also appears in the dialog combo box. If the descriptive text itself contains blanks, the text must be enclosed in quotation marks.

Example of tplinfo.txt file:

```
din.tpl "DIN (Deutsche Industrie Norm)"
kreischer.tpl Kreischer
s&h.tpl Spindler&Hoyer
kodak.tpl Kodak
liebmann.tpl Liebmann
lightnin.tpl Lightning
ofr.tpl OFR
optolyth.tpl Optolyth
```

## 23.7 ISO Element Drawing

Element drawings in accordance to the ISO 10110 standard can be generated from the lens prescription data. Such drawings are useful when a lens design is prepared for fabrication. The tolerances used in element drawings are taken from the previously entered or calculated tolerances.

Element drawings are created by the command

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ELE [ sk   ? ]	Element drawing according to ISO 10110, starting from surface sk.
	Drawing items are taken from prescription data and (where available)
	from tolerance data. The optional question mark invokes a dialog
	box (see Fig. 23.7) for editing drawing items. The drawing can be
	immediately printed/plotted using the redirection symbol, for example
	ELE $s3 > plt$ .

One drawing is generated for each element. Multiple elements must be printed separately. Single lenses or cemented doublets can be drawn. Only centered (axially symmetric) elements are drawn correctly. Tilts or decenter in an element are not reproduced.



Figure 23.7: ISO element drawing dialog box for editing element drawing indications (left) and corresponding sample output (right). The dialog box is invoked from the command line by the command ELE ?.

The dialog box as shown in Fig. 23.7 is the central focus for editing and controlling the appearance of the element drawings. Changes take effect immediately and can be viewed interactively in the associated preview window, which remains open as long as the ISO element drawing dialog box is opened.

Data entry in the dialog box is grouped in six tabbed sections. The first three tabs belong to the first surface, the material and the last surface of a lens. Title information can be entered independently for each lens in the sixth tab. The fourth and fifth tab are reserved for cemented doublets and are activated only when doublet drawing is required (selected from the menu in the upper right corner of the dialog).

Tolerances in the ISO element drawing dialog are automatically taken from the current tolerance data if specified in the tolerance spreadsheet editor (see chapter 22), however, they can always be overwritten by manually entered tolerances.

The tolerances from the tolerance analysis are adapted only once when the corresponding fields in the lens drawing are still undefined. The tolerances in the element drawings are totally independent from the tolerance spreadsheet editor, that is, if you change individual tolerances later, the ELE drawings are not updated. However, you can do this manually by the command:

#### ELE TOLUPD

which updates (synchronizes) changed tolerances in the element drawings.

Element drawing data is retained in the lens file if the appropriate check box "*Save element drawing data with the prescription data*" in the dialog as shown in Fig. 23.7 is checked. Otherwise, element drawing data are lost on program exit or when a new optical system is restored (loaded).

The following description gives a concise overview about the meaning of all data entry fields in the ISO element drawing dialog box. It does not replace a detailed study of the ISO 10110, Parts 1-11, specifications.

- **Radius:** The radius of curvature is taken from the prescription data and cannot be changed in the element drawing dialog. In order to produce manufacturing ready drawings, it is assumed that the radii have been fitted to test plates (see section 23.5). Concave surfaces are denoted by "CC" and convex surfaces are denoted by "CX".
- **Clear Diameter:** Initially the clear diameter is taken from the prescription data and constitutes the effective optical diameter which is required by all defined ray bundles. Note that the clear diameter can be automatically determined by the command SET MHT (set maximum heights). The clear diameter can always be overwritten by the user.
- **Mech. Diameter:** The outside diameter of the element can be specified with a  $\pm$  tolerance. The diameter must be greater or equal to the clear diameter.
  - Chamfer: Minimum and maximum permissible widths of the protective chamfers. Pertains to all edges and corners that are not explicitly specified.
  - **Coating:** Coatings may be specified in a text field. No predefined form is given as coating specifications typically require separate specification documents. Usually, the coating indication contains a reference to the specification document.
  - **Surface Form:** Definition and specification of the surface form is given in detail in ISO 10110, Part 5. Surface form deviation is *"the distance between the optical surface under test and the nominal theo-retical surface, measured perpendicular to the theoretical surface, which shall be nominally parallel to the surface under test."*

Surface form deviation is indicated in fringe spacing (one-half the wavelength of light at 546nm) in one of the three forms:

3/A(B/C) 3/A(B/C) RMSx ; D, where x is either t, i or a. 3/ - RMSx ; D

where

A is the maximum permissible sagitta error in fringes,

**B** is the maximum permissible value of irregularity expressed in fringe spacings,

C is the maximum permissible rotationally symmetric irregularity expressed in fringe spacings, D is the maximum permissible value for rms residual deviation. Only RMSi values can be specified in the dialog box.

**Centering:** Indicates the maximum permissible tilt angle in minutes of arc.

Imperfections: Specifies surface imperfections (scratches, pits and coating blemishes) in the form

5/NxA; C N'xA'; L N"xA"; E A""

where

NxA is the number and size of general surface imperfections,
C N'xA' indicates coating blemishes, where N' is the number of allowed blemishes and A' indicates the grade number,

L N"xA" indicates the long scratch specification with N" being the number of allowed long scratches (>2mm) and A" is the maximum with of the scratches,

**E** A''' is the edge chip specification where A''' specifies the maximum permissible extent of a chip from the physical edge of the surface.

- Material: The material (glass) name is taken from the prescription data and cannot be edited.
  - **nd:** The index of refraction at the d-line (587.6nm). Only the tolerance on refractive index can be specified. The default value is 0.001.
  - Vd: The Abbe number at the d-line (587.6nm). Only the tolerance on Abbe number can be specified. The default value is 0.8%.
  - **Stress Birefringence:** It is specified in terms of optical path difference, expressed in nm/cm. The default value is 10nm/cm.
- **Bubbles and Inclusions:** The specification is indicated by 1/ NxA, where N is the allowed number of bubbles and inclusions and A is a grade number. See ISO 10110 Part 3 for further reading.
  - Striae and Inhomogeneity: The specification is indicated by 2/ A;B, where A is the inhomogeneity and B is the striae class. Inhomogeneity is characterized by the maximum permissible variation in refractive index, given in 10<sup>-6</sup> units. Striae is defined in five classes where classes 1-4 are related to a density of striae. Class 5 is virtually free of striae and requires further information in a note. See ISO 10110 Part 4 for further reading.
- Thickness: The tolerance on axial thickness.
  - **Mirror Thickness:** This field is only active on mirror surfaces. The mirror thickness is the center thickness to the back surface of a first-surface mirror. In the command line, this value is specified by the THM command.
    - **Part:** The element can be identified by a part name. Even though it is possible to enter a part name for every surface, only the part name of the leftmost surface of the element/doublet appears on the drawing.
- Part No.: A number identifying the element. The field is limited to 64 characters.
- Revision: Tracks version changes. The field is limited to 64 characters.
- **Remarks:** A text field limited to 64 characters for entering additional notes.

### 23.8 CAM Calculation

The CAM option provides a table of parameters for constructing a precise relationship between movable parts (lenses or groups of lenses). This option is preferably used in constructing the cam for a mechanically compensated zoom lens, however, it is not restricted to calculate axial separations but allows *any* lens parameter to be included in the calculation. Thus, in OpTaliX CAM may also be used for calculating relationships between tilt and decenter parameters (for example in scanning systems) or any other exotic combination of description parameters.

CAM generates cam data by optimizing the optical system at each step of the cam. This is done by successive passes through the optimization option incrementing the linear variable (stepping) parameter **STE** before each pass.

The CAM option does not primarily require a zoomed system, or that the system is 'dezoomed' prior to calculating cam tables. CAM mode is universally available for both zoomed and non-zoomed (fixed focus) systems.

In order to facilitate this capability, OpTaliX provides two completely independent data areas to hold optimization variables, targets and constraints, which do not interfere. That way, 'normal' optimization and CAM calculation can be performed independently in the same setup.

Two modes of operation are provided, a 'normal' zoom mode and a CAM mode. Switching between those two modes is accomplished by the commands "CAM Y" and "CAM N".

In the description to follow we will concentrate on the most often required case of mechanically compensated zoom lenses, that is, the computation of a table of axial separations between moved groups.

In a zoomed system, simply switch to CAM mode, define a second optimization set and perform CAM calculation. Then the user may switch back to normal zoom/multi-configuration mode and continue optimization or analysis of the zoomed system. OpTaliX saves both optimization sets with the prescription data. This allows continuation of 'normal' zoom optimization/analysis and/or CAM calculation from saved and restored systems.

Also note that due to the close relationship of CAM calculation and optimization settings, menu items to edit CAM parameters are found both in the *Optimization* and *Manufacturing* main menus.

When switching to CAM mode in a zoomed system, the program temporarily converts the system to a non-zoomed system (without losing the zoom data!) and calculates the cam. The previous zoomed state can always be restored by the "CAM N" command.

CAM Y N zk RUN [XLS file.xls]	Switch between CAM mode (Y) and normal zoom mode (N). Automatically dezooms a system to position 1. Specify zk to start CAM calculation from any other position zk. If in CAM mode, CAM calculation can be initiated by the RUN parameter. The XLS option exports the cam table to an Excel file. See also the notes on creating an Excel file (page 502).	
	Ine. See also the notes on creating an Excel file (page 502).Examples:CAM Y! switch to CAM mode starting with position 1,CAM z2! switch to CAM mode starting with position 2,CAM RUN! execute CAM calculation,CAM N! switch back to normal zoom mode.CAM RUN XLS c:\my_data.xls! execute CAMand export data to Excel file.	
	continued on next page	

#### Commands:

continued from previous page	
STE sk param	
or CAM STE sk param	Designates the separation or parameter to be stepped linearly. If only a surface qualifier is specified, separation of that sur- face is assumed. That is, sk is implicitly understood as "THI sk". It is, however, possible to specify <i>any</i> prescription pa- rameter, which is specified in the param string.
	For example,STE s5! steps separation 5 (THI s5) linearly,STE ADE s7! steps tilt about X-axis on surface 7(ADE s7) linearly,STE 'ADE s7'! as above but param provided asstring.
INC step_size	
or CAM INC step_size	Size of step to be taken in the separation or parameter target.
LIM max_value	
or CAM LIM max_value	Stop the CAM calculation when the value of the stepped sepa- ration/parameter (given by STE) exceeds this value.
CAM OUT param_string110	Designates up to 10 parameters for which values are listed. The parameter definitions must be provided as strings, that is they must be enclosed in quotes. Parameter strings must be separated by at least one blank character. Parameter strings do not (yet) accept lens database items and arithmetic expres- sions. Example: CAM OUT 'thi s5' 'thi s10' 'efl' 'oal'
BAS offset	
or CAM BAS offset	Designates a constant value to be added to each of the listed parameters. Allows matching of table to reference points in the mechanical design.
LIS CAM	List CAM parameter and associated CAM optimization vari- ables and constraints.
EDI CAM	Edit CAM parameter and associated CAM optimization vari- ables and constraints in a dialog box.

Upon exit from a cam calculation in the CAM mode, the system is left in the configuration of the last cam step so that a continued run (with different parameters) may be made if desired. If the system is later switched to normal zoom mode (see CAM N command), the optical system is restored at zoom position 1.

### Example:

The CAM calculations performed in this example are based on the design CAM\_Example.otx found in the <code>\optalix\examples</code> optimization directory. In this design, thicknesses 5, 10 and 15

are variable to accomplish the movement of the groups. Thickness 5 will be linearly stepped through the allowable movement range (1mm - 50mm). The remaining thicknesses 10, 15 are optimized to fulfil a constant focus on the optical axis and a constant overall length (OAL).

We enter the CAM mode,

CAM Y

and define the linear stepping parameter

STE	THI s5	! Step thickness on surface 5
INC	2.0	! Increment for surface 5
LIM	50.0	! Maximum value of surface 5

The variables and targets/constraints for CAM calculation are defined in the same way as for normal optimization. Variables can be edited in a dialog (use VAR ? command) or directly from the command line:

```
VAR s10 THI
VAR s15 THI
```

The targets/constraints definition for CAM calculation is short and sweet:

spd f1 0 ! Minimize spot diameter at field 1 (axis), oal = 121.5 ! Maintain overall length (OAL).

Finally we need to define the parameters to be listed. These are the thicknesses 10 and 15. In addition we want to monitor focal length (EFL) and the overall length (OAL).

CAM OUT 'thi s5' 'thi s10' 'efl' 'oal' 'spd f1'

Note that the parameters to be listed must be given as strings (that is enclosed in apostrophes) and parameter strings must be separated by at least one blank character.

Here is a summary of the whole story, obtained by the LIS CAM command:

CAM CALCULATION PARAMETERS: Linear stepping parameter Stepping increment Maximum of stepped parameter	(STE) (INC) (LIM)	: THI : :	s5 2.00000 50.00000
List Parameter	Off	Iset	
1 : INI 510	0.0	0000	
2 : IHI 515	0.0	1000	
3 : EFL	0.0	0000	
4 : OAL	0.0	0000	
5 : SPD F1	0.0	000	
CAM VARIABLES :			
S10 THI			
S15 THI			
CAM TARGETS AND CONSTRAINTS : spd f1 0 oal = 121.5			

The cam calculation is initiated by the command CAM RUN:

CAM CALCULATION FILE = CAM\_Example.otx THI S5 THI S10 THI S15 EFL OAL SPD F1

1	1.00000	56.47201	1.12499	5.90331	121.50000	0.00367
2	3.00000	54.37153	1.22547	6.25214	121.50000	0.00354
3	5.00000	52.26517	1.33183	6.63267	121.50000	0.00343
4	7.00000	50.15151	1.44549	7.04912	121.50000	0.00338
5	9.00000	48.03185	1.56515	7.50546	121.50000	0.00330
6	11.00000	45.90509	1.69191	8.00707	121.50000	0.00324
7	13.00000	43.76938	1.82762	8.56059	121.50000	0.00325
8	15.00000	41.62445	1.97255	9.17309	121.50000	0.00333
9	17.00000	39.46936	2.12764	9.85319	121.50000	0.00348
10	19.00000	37.30302	2.29398	10.61110	121.50000	0.00373
11	21.00000	35.12420	2.47280	11.45900	121.50000	0.00411
12	23.00000	32.93149	2.66551	12.41154	121.50000	0.00463
13	25.00000	30.72328	2.87372	13.48641	121.50000	0.00529
14	27.00000	28.49768	3.09932	14.70510	121.50000	0.00609
15	29.00000	26.25255	3.34445	16.09395	121.50000	0.00700
16	31.00000	23.98536	3.61164	17.68545	121.50000	0.00801
17	33.00000	21.69320	3.90380	19.51995	121.50000	0.00913
18	35.00000	19.37267	4.22433	21.64797	121.50000	0.01033
19	37.00000	17.01982	4.57718	24.13323	121.50000	0.01159
20	39.00000	14.63009	4.96691	27.05663	121.50000	0.01284
21	41.00000	12.19831	5.39869	30.52153	121.50000	0.01397
22	43.00000	9.71879	5.87821	34.66022	121.50000	0.01478
23	45.00000	7.18589	6.41111	39.64128	121.50000	0.01493
24	47.00000	4.59570	7.00130	45.67467	121.50000	0.01383
25	49.00000	1.95113	7.64587	53.00207	121.50000	0.01075

INFORMATION: The system has been left at the last step in the CAM Enter "CAM N" to restore all zoom positions (Zoom systems only).

Short form	Manufacturer
app	Applied Optics
bm	B&M Optik
bef	Befort
ber	Bern Optics
br1	Brighten Optics, Shop 1
br2	Brighten Optics, Shop 2
br3	Brighten Optics, Shop 3
coa	Coastal Optical Systems
com	Computer Optics Inc.
con	Continental Optical Corp
ddo	DD-optik
din	DIN (Deutsche Industrie Norm)
gos	GOST Russian testplates
har	Harold Johnson Optical Lab.
ii-	II-IV Incorporated
ian	Janos
ilw	JLWood Optical Systems
kod	Kodak
kre	Kreischer
lig	Lightning
lie	Liebmann
lin	Linos
mel	Melles Griot
mod	Model Optics
med	MediVision
nee	Neeb Ontik
new	Newport
oci	OCI (Optical Components Inc.)
ofr	OFR (Optics for Research)
ogf	OGF (Optico Glass Fabrication)
opt	Optimax
opl	opl Optolyth
pog	Praezisionsoptik Gera
pro	PRO (Pacific Rim Optical)
rmi	Rocky Mountain Instruments
rod	Rodenstock
sil	Sill Tools
spe	Special Optics
spc	Spectros
swi	ŚwissOptik
tel	Telic Optics
tro	Tropel Corp.
tuc	Tucson Optical Research Corp.
tow	Tower

Table 23.1: Available test plate lists and corresponding 3-letter short forms.

# **Glass Manager**

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OpTaliX contains a number of auxiliary tools to select, view and analyze optical properties of glasses.

### 24.1 Use of Glass Catalogs

This section describes the use of glass catalogs. Typically, one or multiple glass catalogs can be loaded for a particular optical system. The following commands support this feature:

	Load glass catalogues, designated by a sequence of catalogue names, e.g.
LOAD GCAT cat1 cat2 cat3	load gcat schott hoya oha
	would load the glass catalogs from Schott, Hoya and Ohara. Only the first three characters are significant.
LOAD GCAT ALL   ?	As above, loads glass catalogues. The parameter ALL loads all glass catalogs that are available in $OpTaliX$ . The question mark "?" invokes a dialog box for interactive selection of catalogues.
LIS GCAT	Lists the currently loaded glass catalogues in the text output window.

Alternatively, interactive selection of glass catalogues is accomplished by from the main menu

*Glass Manager* --> *Select Glass Catalogs* 

A dialog box is invoked which allows selection of particular glass catalogs or all glass catalogs that are available in OpTaliX (see Fig. 24.1).

### 24.2 Glass Map

The glass map is a diagram of index of refraction versus Abbe number  $\nu$  or versus dispersion  $n_F - n_C$  as provided by most glass manufacturers. The collection of glass catalogues is selectable by the command LOAD GCAT ?.



Figure 24.1: Selection of particular glass catalogs using the command "LOAD GCAT ?" (without quotes).

NNU	Plot glass map, index of refraction vs. Abbe number
NFNC [?]	Plot partial dispersion diagram. Use the optional "?" pa-
	rameter to invoke a dialog for selecting glass catalogues
	and diagram options. See also sect. 24.3 below.

# 24.3 Partial Dispersion Plots

The partial dispersion plots are invoked by the NFNC command and show the deviation of the glass dispersion from the Abbe normal line (defined as a straight line connecting the Schott glasses K7 and F2). The selectable partial dispersions are  $P_{g,F}$ ,  $P_{C,s}$ , two artificial partial dispersions for the spectral regions  $1 - 2\mu m$  and  $3 - 5\mu m$ , and a plot of the partial dispersions  $P_{g,F} - P_{d,C}$ . For the latter, a similar plot is available using the Buchdahl coefficients  $\eta_1, \eta_2$ .

# 24.4 Athermal Map

The athermal map plots chromatic dispersive power versus thermal dispersive power, see Fig. 24.5. This is a useful tool for finding optical systems corrected for both chromatic aberrations and focus shift over temperature. See also section 24.5 for a more analytical approach to this subject.

For each material, chromatic dispersive power  $\omega$  and thermal power  $\psi$  can be computed as

$$\omega = -\frac{(\partial n/\partial \lambda)\Delta\lambda}{n-1}$$
(24.1)

$$\psi = \frac{\partial n/\partial T}{n-1} - \alpha \tag{24.2}$$



Figure 24.2: Glass maps, shown for Schott glasses. Left: index of refraction vs. Abbe number, right: index of refraction vs. dispersion  $n_F - n_C$ .

where  $\alpha$  is the linear expansion coefficient. Note that the chromatic dispersive power  $\omega$  is proportional to  $1/\nu$ , where  $\nu$  is the Abbe number as defined in Eq. 13.14 (page 223). For the sake of simplicity, we consider a thin-lens doublet (i.e. two materials) only, which we want to achromatize (zero chromatic dispersive power) and athermalize (zero thermal power). This requires the solution of three linear equations,

$$\Phi = \Phi_1 + \Phi_2 = 1 \tag{24.3}$$

$$\Delta \Phi = \omega_1 \cdot \Phi_1 + \omega_2 \cdot \Phi_2 \tag{24.4}$$

$$\frac{d\Phi}{dT} = \psi_1 \cdot \Phi_1 + \psi_2 \cdot \Phi_2 \tag{24.5}$$

Referring to Fig. 24.5, this means that the two materials should lie on a straight line O-L intersecting the origin O in the thermal map. If no such material combination can be found, in particular when materials must transmit in a non-visible wavelength range (e.g. infrared glasses), three materials must be combined to accomplish the desired effect. For further reading see Tamagawa et.al. [55],[56].

#### Notes:

The athermal map does NOT take into account thermal effects of the housing structure (i.e. changes of air spaces under temperature), lens thicknesses and higher order ray aberrations. Therefore, in real systems, the athermal map can only be used as a guideline for selecting materials suitable for athermalization.

The following section 24.5 describes a method to include effects of housing expansion, at least in the paraxial domain.

# 24.5 Athermal Glass Selection

Tamagawa et.al. have devised a numerical method for athermalizing optical systems by combining optical materials with suitable lens powers and simultaneously fulfilling the achromaticity condition [54], [55], [56]. The method is based on determining both thermal and dispersive powers and calculating the corresponding lens powers, including the effects of thermal housing expansion.

Because it is difficult to find pairs of two glasses that lie on a straight line going through the origin of the athermal glass map (Fig. 24.5), accomplishing an athermal doublet is unlikely, albeit not



Figure 24.3: Partial dispersion plots, shown with Schott glasses. Left: index of refraction vs.  $P_{g,F}$ , right: index of refraction vs.  $P_{C,s}$ .

impossible. The following treatment focusses on a combination of three materials (triplet) which gives more flexibility and always allows to find suitable glass combinations for a given application.

With three glasses, we have three equations to be simultaneously fulfilled:

$$\Phi = \Phi_1 + \Phi_2 + \Phi_3 = 1 \tag{24.6}$$

$$\Delta \Phi = \omega_1 \cdot \Phi_1 + \omega_2 \cdot \Phi_2 + \omega_3 \cdot \Phi_3 \tag{24.7}$$

$$\frac{d\Phi}{dT} = \psi_1 \cdot \Phi_1 + \psi_2 \cdot \Phi_2 + \psi_3 \cdot \Phi_3 \tag{24.8}$$

These equations can be expressed in matrix form,

$$\begin{bmatrix} \Phi_1 \\ \Phi_2 \\ \Phi_3 \end{bmatrix} \cdot \begin{bmatrix} 1 & 1 & 1 \\ \omega_1 & \omega_2 & \omega_3 \\ \psi_1 & \psi_2 & \psi_3 \end{bmatrix} = \begin{bmatrix} \Phi \\ 0 \\ -\alpha_h l\Phi \end{bmatrix}$$
(24.9)

The thermal expansion of the housing is considered by  $-\alpha_h l\Phi$  where  $\alpha_h$  is the linear expansion coefficient of the housing material and l is the length of the housing. The individual lens powers are then obtained by

$$\begin{bmatrix} \Phi_1 \\ \Phi_2 \\ \Phi_3 \end{bmatrix} = M^{-1} \begin{bmatrix} \Phi \\ 0 \\ -\alpha_h l\Phi \end{bmatrix}$$
(24.10)

It is important to note that the above equations refer to the paraxial domain. Solutions of Eq. 24.10 do not necessarily result in systems with good aberration correction. It is therefore advisable to search for glass combinations with minimum individual lens powers  $\Phi_1, \Phi_2$  and  $\Phi_3$ .

#### **Command Input:**

ATH3	Find three-glass combinations for athermal and achromatic correction
	in the paraxial domain.



Figure 24.4: Partial dispersion plots with Buchdahl coefficients  $\eta_1, \eta_2$ , shown for Schott glasses.

# 24.6 Glass Selection for Thin-Lens Apochromats

This option is intended as an aid to selecting glass combinations, which are suitable for achieving apochromatic colour correction. Combinations of two and three glasses are supported. In finding such combinations, the program compares the dispersion properties of all glasses against a *base glass* and prints the required powers of the individual lenses.

The comparisons are based on Buchdahl's simplified equations for modeling dispersion by introducing a change in variables from wavelength  $\lambda$  to a chromatic coordinate  $\omega$ . It is defined as

$$\omega = \frac{\lambda - \lambda_0}{1 + \frac{5}{2} \left(\lambda - \lambda_0\right)} \tag{24.11}$$

where  $\lambda_0$  is the reference wavelength.

Using the chromatic coordinate, the index at any wavelength is expressed by the power series

$$n = n_0 + \nu_1 \omega + \nu_2 \omega^2 + \dots + \nu_i \omega^i$$
(24.12)

where  $n_0$  is the index at the reference wavelength  $\lambda_0$  and the quantities  $\nu_1, \nu_2, ...$ , characterize the dispersion of the glass. This Taylor series converges very rapidly. The dispersive properties of glass are modelled with sufficient accuracy in the visible range (400-700nm) by a quadratic equation, and in the range 400 - 1000nm by a cubic equation.

It is important to note, that the above equations, if applied to real glasses and optical systems, are only valid in the paraxial domain. However, it may turn out that certain combinations will not perform as expected. In almost all cases, this is due to higher order monochromatic and chromatic spherical aberration, which is not covered by paraxial quantities.

#### 24.6.1 Two-Glass Apochromats

APO2 [ base_glass   ? ]	Find two-glass combinations forming apochromatic cor-
	rection in the paraxial domain.



Figure 24.5: Athermal map, plotting chromatic dispersive power vs. thermal power for Schott glasses in the visible spectral range.

#### **Example:**

For a given base glass, the command APO2 selects glass combinations, where the ratio of the dispersion coefficients is as identical as possible to another glass.

The output gives a list of matching glasses (including their equivalent name) and the lens powers for a doublet of power = 1. The last column shows the expected rms-error of the longitudinal chromatic aberration (secondary spectrum) in the *paraxial* domain. Promising combinations are those with small lens powers (Phi1, Phi2) and small rms-error. However, even if the rms-error is small, high lens powers indicate large amounts of higher order chromatic aberrations (spherochromatism).

```
Glass dispersion coefficients based on Buchdahl chromatic coordinates :
Baseglass : KZFSN4
        : -0.14080
: 0.04012
 Eta_1
 Eta_2
 Ref.wavelength :
                    0.5500 micron
Glass
              Equiv.Glass
                              Phi1
                                       Phi2
                                                   RMS
SCH:LLF1
              N-LLF1
                           -30.308
                                    31.308
                                                0.3855
SCH:N-BAF3
                                    20.172
              BAM3
                           -19.172
                                                0.2716
SCH:N-BAF10
              S-BAH10
                           -15.614
                                     16.614
                                                0.0964
SCH:N-BAF51
              N-BAF51
                           -64.353
                                      65.353
                                                0.9895
SCH:N-KF9
              N-KF9
                            -6.107
                                      7.107
                                                0.0631
SCH:N-KZFS4
              N-KZFS4
                          -206.546 207.546
                                                0.7215
SCH:N-KZFS11
              N-KZFS11
                           23.824
                                    -22.824
                                                0.0012
SCH:N-LAF2
              N-LAF2
                           -75.176
                                      76.176
                                                0.9451
. . . . . . .
```

#### 24.6.2 Three-Glass Apochromats

APO3 [ base_glass   ? ]	Find three-glass combinations forming apochromatic
	correction in the paraxial domain.

The following output is an example list for the base glass KZFSN4 from Schott:

```
Glass dispersion coefficients based on Buchdahl chromatic coordinates :
Baseglass : KZFSN4
Eta_1
       : -0.14080
: 0.04012
Eta_2
Ref.wavelength : 0.5500 micron
                                                Phi1
                                                          Phi2
                                                                   Phi3
Glass1
              Glass2
                            Glass3
SCH:KZFSN4
                             SCH:N-FK51
                                               -2.906
                                                          1.238
                                                                   2.669
              SCH:F2
                                                                   2.313
                                               -2.387
SCH:KZFSN4
              SCH:F2
                            SCH:N-FK56
                                                          1.074
SCH:KZFSN4
             SCH:F2
                            SCH:N-PK52
                                               -2.913
                                                         1.171
                                                                   2.742
SCH:KZFSN4
            SCH:F5
                            SCH:N-FK56
                                               -2.568
                                                         1.294
                                                                   2.274
                           SCH:N-FK56
            SCH:LAFN7
                                               -2.533
SCH:KZFSN4
                                                          1.105
                                                                   2.428
SCH:KZFSN4
              SCH:LASFN9
                             SCH:N-FK51
                                               -2.458
                                                          0.756
                                                                   2.701
SCH:KZFSN4
              SCH:LASFN9
                             SCH:N-FK56
                                               -1.993
                                                         0.655
                                                                   2.337
                           SCH:N-PK52
                                               -2.489
                                                       0.715
                                                                   2.774
SCH:KZFSN4
            SCH:LASFN9
SCH:KZFSN4
            SCH:SF1
                             SCH:N-FK51
                                               -2.359
                                                         0.613
                                                                   2.747
. . . . . . .
```

# 24.7 Gradient Index Profile

The profile of gradient index glasses shows the index of refraction as a function of the local zcoordinate. Currently, this plot is only available for pre-stored gradient index glasses with *axial* gradient. The plots are shown at the selected wavelengths.



Figure 24.6: Gradient index profile, shown for five wavelengths.

# 24.8 View and Edit Glass Catalogues

	Invokes a spreadsheet containing glass data stored in the glass cat- alogues. The optional parameter cat_name is a three-character string designating the catalogue. The following catalogues are available:		
	cat_name	Glass manufacturer	
	SCH	Schott	
	SCO	Old Schott	
	OHA	Ohara	
	НОҮ	Ноуа	
	COR	Corning	
GCAT [cat name]	SUM	Sumita	
	CAR	Cargille liquids	
	LPT	LightPath Gradium	
	SPE	Specials catalogue (infrared, plastic,	
		etc.)	
	HIK	Hikari	
	CHI	Chinese catalogue	
	MLT	Melts (user defined glasses)	
	Examples:		
	gcat		
	gcat sch		

Only the melts catalogue (MLT) may be edited and saved whereas the data of all other catalogues can only be viewed. This is mandatory in order to preserve data integrity of glass catalogues during later updates.

<sup>s </sup> Glass Cata	logue Editor	Schott						_ 🗆 ×
Schott		Glass Name	Equiv.Name	Index (d)	Nue (d)	Coef. 1	Coef. 2	Coef. 3 🔺
	F2	F2	F2	1.620037	36.35	1.3453336	0.20907318	0.93735716
Uld Schott	F5	F5	F5	1.603417	38.01	1.3104463	0.19603426	0.96612977
Ohara	K7	K7	K7	1.511119	60.38	1.1273555	0.12441230	0.82710053
Houa	K10	K10	K10	1.501369	56.39	1.1568708	0.64262544E-01	0.87237614
	LAFN7	LAFN7	LAFN7	1.749498	34.94	1.6684262	0.29851280	1.0774376
Corning	LAKN13	LAKN13	LAKN13	1.693499	53.31	1.2579237	0.55340286	1.0633574
Sumita	LASFN9	LASFN9	LASFN9	1.850250	32.16	1.9788819	0.32043530	1.9290075
Hikori	SF1	SF1	SF1	1.717355	29.50	1.5591292	0.28424629	0.96884293
HIKdii	SF10	SF10	SF10	1.728245	28.40	1.6162598	0.25922933	1.0776232
Cargille	SF11	SF11	SF11	1.784714	25.75	1.7384840	0.31116897	1.1749087
LightPath	SF14	SF14	SF14	1.761814	26.52	1.6918254	0.28591993	1.1259515
	SF15	SF15	SF15	1.698947	30.06	1.5392593	0.24762093	1.0381641
Special	SF2	SF2	SF2	1.647685	33.83	1.4030182	0.23176750	0.93905655
	CEA	SF4	SF4	1 755196	27 57	1 6195783	N 33949319	1.0256693



The meaning of the columns is as follows:

Glass Name	The manufacturers glass name
Equiv.Name	Glass name of an equivalent glass. That is its optical properties are
	very similar. This can also be a glass from an other manufacturer.
Index(d)	Index of refraction at d-line
Nue (d)	Abbe number $\nu_d$
Coef. 1-6	Dispersion coefficients. The type of dispersion formula is defined
	in the Column "Eq".
	Type of dispersion formula
Fa	0 = Old Schott formula, see Eq. 13.1 page 221.
Lq.	1 = Sellmeier formula, see Eq. 13.2 page 221.
	2 = Herzberger formula, see Eq. 13.8 page 222.
L-min	minimum wavelength in $\mu m$ for which the dispersion coefficients
	are valid.
L-max	maximum wavelength in $\mu m$ for which the dispersion coefficients
	are valid.
D0	
D1	
D2	Temperature coefficients $dn/dT$ of index of refraction according
E1	to Eq. 13.2.
E2	1
	The much coefficient of expression in $10^{-6}$ units
	I hermal coefficient of expansion in $10^{\circ}$ units.
Rho	Specific gravity $\rho$ in $g/cm^3$ .
RII	Thickness in mm for which internal transmission data are defined.
2500 - 250	Internal transmission (excluding reflection losses) for a glass plate
	of thickness R'fI at the wavelength (in nm) given in the column
	heading.

# 24.9 Melt Glasses

Manufactured optical glass and other materials as well vary slightly in refractive index from batch to batch as compared to the nominal or catalogue value. Typical tolerances for optical glass as supplied without any other specification are  $n_d \pm 0.001$  and  $\nu_d \pm 0.8\%$ .

For critical applications such as long-focal-length high-resolution types, such (standard) tolerances are not sufficient and analysis with the exact measured refractive index data must be performed. To aid this process, glass manufacturers generally supply melt data sheets for each batch of glass, which allows adjustment of the values of radii, lens thicknesses or air spaces. Typically, the data is provided by the glass manufacturer at the wavelengths of a few selected spectral lines and some sort of fitting is required to obtain refractive index data at the wavelengths for which the optical system is designed. The interpolation uses the Sellmeier equation as described in equation 13.2.

In order to use measured melt data, a new glass must be created on the basis of the manufacturer's melt data sheet and then added to the (melt) glass catalogue. Once created, the melt glass can be used like any ordinary catalogue glass.

This method is very general and can be used not only for melt glasses (i.e. glasses which deviate only slightly from a pre-stored catalogue glass) but also for creating entirely new glasses. Any feasible wavelength range may be entered, thus also "infrared" glasses or "UV" glasses may be created this way. It is, however, important to note that this scheme only applies for *homogeneous* glasses/materials. Inhomogeneous glasses such as gradient index cannot be created with this option. **Commands:** 

MELT [? fil	Create a melt glass from a set of discrete wavelength/index of pairs. Interpolation to Sellmeier coefficients is performed and melt glass is then added to the "melts" catalogue. For comm line input, the wavelength/index data pairs must be stored in ASCII-file with extension ".ind". The melt glass file form is described in section 32.8. When used with the "?" option dialog box is invoked for interactive editing.
melt_file_name]	Examples: melt fil c:\optix\glasses\my_melt.ind Fits index data contained in a file. melt ? Invokes dialog box for melt data editing

#### **Dialog based Creation of Melt Glasses:**

A particulary convenient method of creating and fitting melt glasses is using the dialog box. It is invoked by the command "MELT ?" or from the main menu *Glass Manager*  $\rightarrow$  *Create Melt Glass*.



Figure 24.8: Dialog box for entering, fitting and creating melt glasses and new glasses respectively.

Two types of index data may be entered, either

- from the Schott melt data sheet (check the "*Schott melt data sheet*" radio button). The data must be entered manually into the dialog fields,
- or as pairs of wavelength/index data (check the "*Measured index data*" radio button. This data can be entered manually or can be restored from an ".ind" file, which should be preferably stored in the \optix\melts\ directory (but may be any other).

Using the example dialog shown in Fig. 24.8, the steps to creating a melt glass are

1. Enter the wavelength/index pairs or load it to the dialog from an ".ind" file in the melts directory (click on the "load indices" button underneath the wavelength/index spreadsheet). Check those wavelengths, which shall be included into the fit. A maximum of 100 wavelength/index data pairs may be entered.

- 2. Select the formula to which the data shall be fitted. Currently, the old Schott equation (Eq. 13.1) and the Sellmeier equation (Eq. 13.2) are selectable.
- 3. Fit the data according to selected formula (click the "fit coeffs." button). The coefficients are then displayed in the rightmost table and are also reported (along with the accuracy of the fit) in the text window.
- 4. Enter a name for the new melt glass. A unique name (maximum 10 characters) must be given to identify the melt glass and distinguish it from the other catalogue glasses.
- 5. Select (or enter directly) a "base" glass name, from which other glass properties (such as internal transmission, dn/dT, CTE, specific gravity, etc.) are taken and are also assigned to the new melt glass. In this way the melt glass possesses all properties of the base glass and behaves identically to the base glass (except index of refraction) for all subsequent analyses. Thus, analyses on transmission, thermal expansion, weight, etc. produce the same results for melt glass and base glass.
- 6. Add the fitted glass to the melts catalogue (press the "Add" button).
- 7. Close the dialog box.

# **Printing and Plotting**

Throughout this section, the term "printing" is understood as printing text to the printer, i.e. all text and analysis output, which normally appears in the "text window" on the screen. The term "plotting" is denoted as "printing" graphics to the printer using the Windows print manager. By default, all graphics and analysis output is directed to screen windows. To perform printing or plotting, the output device must be changed. Once an output unit is changed, all subsequent outputs are directed to the chosen device. To display the graphics and/or text output on the screen again, the corresponding output must be switched back to the screen. This concept works like a light switch, which is turned on and off. The currently selected output device (graphics or text) is displayed in the status bar of the main window as indicated in Fig. 25.1.



Figure 25.1: Print status shown in the status bar at the bottom of the main window.

In order to print/plot from the command line, you must switch the output devices manually as described in the following sections. From the GUI, switching output devices is done automatically in the background.

# 25.1 Printing and Plotting from the Command Line

out prn   t   file	Direct text output to the default printer (prn) or the ter-
file_name	minal/screen (t). Text output can be written to a file
	with the command out fil file_name. See exam-
	ples below.
gra prn plt t file	Direct graphics output to the printer (prn), plotter
	(plt), screen or text output window (t), or to a file
	(fil).
	continued on next page

# 25

continued from previous page	
bmpx pixels_horiz	Number of horizontal pixels in writing bitmaps (BMP, PCX). See sect. 25.2.2 for an example. The default width is 640 pixels.
bmpy pixels_vert	Number of vertical pixels for writing bitmaps (BMP, PCX). See sect. 25.2.2 for an example. The default height is 480 pixels.

For example, the following commands direct text output to the printer, a file or to the to the screen (text output window):

out prn	! output is directed to the default printer (output device is "prn")
out t	! output is directed (back) to the text output window (terminal)
<pre>out fil 'c:\my output.txt'</pre>	! write text output to file "c:\my output.txt".

In a similar way, changing the plot device (i.e. "printing" graphics) is accomplished by:

gra	prn	! graphics output is directed to the default printer(output device is "prn")
gra	t	! graphics output is directed back to the screen.

# **25.2** Printer and Plotter Device Units

The following output devices exist for printing text and plotting graphics:

prn	the default printer	text + graphics
plt	the plotter	graphics only
t	Screen (terminal)	text + graphics
clp	Clipboard	graphics only
file	Text/analysis output to a file	text only
silent	Disables text output (silent operation)	text only
hpgl	HPGL (Hewlett Packard Graphics Language)	graphics only
dxf	Graphics output to AutoCad DXF File	graphics only
eps	Graphics output to Encapsulated Postscript (EPS)	graphics only
wmf	Graphics output to Windows Metafile Format (WMF)	graphics only
cgm	Graphics output to Computer Graphics Metafile (CGM)	graphics only
bmp	Graphics output to Windows Bitmap format (BMP)	graphics only
рсх	Graphics output to Paitbrush file format (PCX)	graphics only
png	Graphics output to Portable Networks Graphics (PNG) format	graphics only
svg	Graphics output to Scalable Vector Graphics (SVG) format	graphics only

The following sections (25.2.1, 25.2.3) describe how printing/plotting is accomplished from the command line. Section 25.3 describes printing/plotting from the graphical user interface (GUI) directly.

### **25.2.1 Printing/Plotting Graphics**

The default graphics output device is the screen. Other graphics output devices may be selected by the following commands:

gra	dxf [file filespec]	! redirect graphics to DXF-File
gra	hpgl [file filespec]	! redirect graphics to HPGL-File
gra	bmp [file filespec]	! redirect graphics to Windows bitmap (BMP) file
gra	prn	! redirect graphics to default printer
gra	plt	! redirect graphics to default printer, synonymous to gra prn
gra	t	! redirect graphics to default screen

Other than for screen, printer and clipboard, graphics are always written to a file and, in this sense, redirecting a graphics output may be understood as "exporting" the contents of a graphics window in the specified format.

For single plots, the graphics may be redirected to the printer/plotter temporarily by using the redirection symbol ">". For example,

fan > plt
vie > plt

redirect the ray-fan or lens layout plot immediately to the corresponding output unit, which is the Printer/Plotter "plt". Note, that the command entries must be separated by at least one single blank character. It is also important to note that the redirection is active only for one particular command, all subsequent commands appear on the previously selected device (usually the screen).

### 25.2.2 Controlling Bitmap Size

The size of graphics exported (printed) to bitmaps (BMP, PCX, Clipboard) can be controlled in two ways:

#### From the GUI:

The size of exported graphics to *raster image files* such as BMP, PCX, as well as to the clipboard corresponds to the size of the graphics window on the screen in pixel. That is, a small graphics window on screen will produce a small raster image file. The file size (and hence the number of pixels in horizontal and vertical direction) increases with increasing screen window size.

#### From the Command Line:

Specify the size of exported graphics by the commands BMPX, BMPY. The following example defines a lens layout plot (VIE command) as a bitmap of 800 pixels wide and 600 pixels high written to the file "c:\my\_graphics.bmp":

```
gra bmp fil c:\my_grahics.bmp
bmpx 800
bmpy 600
vie
gra t
```

Note the logic of exporting graphics: In the command "gra bmp ..." you define an output unit for the graphics (in this case, a file c:\my\_graphics.bmp). Then additional commands can be added to define the property of the graphics such the bitmap size (BMPX, BMPY). Generate the type of graphics and then re-direct the graphics output back to the screen (windows) using the "GRA T" command.

# 25.2.3 Printing Text Output

The default output device for text is the screen (terminal device). Other devices for text output may be selected by the following commands:

out	prn	redirect all subsequent text output to default printer
out	file file_name	redirect all subsequent text output to file_name.
out	t	redirect all subsequent text output to default screen
out	silent	disables text output (silent operation). Use one of the commands
		"out t" or "out prn" to enable text output again.

Once the output is directed to the printer (out prn), all subsequent text outputs will be printed on the default printer until the the text output is switched back to the screen (out t). Text output may be immediately redirected to the printer in a single command with the redirection symbol ">". For example,

lis > prn	! Listing is immediately printed on the default printer.
rsi f1 w1 > prn	! Single ray trace data is redirected to printer
lis > xxx.txt	! output to file xxx.txt

Note, that the command entries must be separated by at least one single blank character! The redirection is active only for one particular command, all subsequent outputs are written to the previously selected device (usually the screen).

# 25.3 Printing/Plotting from the GUI

The previous sections have shown how text/graphics can be printed/plotted from the command line. Whereas this is most useful in macros, for example to automate reports, there is an easier way for printing/plotting text and graphics.

### 25.3.1 Printing Text from the GUI

The entire text displayed in the text window or selected text can be printed.

Printing is then performed by clicking on the printer icon in the main window toolbar (Fig. 25.3).

**Note:** If no text is selected, the contents of the entire window is printed. See also the CLS command for clearing the text window.

### 25.3.2 Printing Graphics from the GUI

Each graphics window has a toolbar to the left. Simply click on the printer icon to print the graphic contents of this window:

### 25.3.3 Examples

#### Send graphics to the clipboard:

gra clp fan gra t

PIM = yes SYM = yes FNO = 2.5	0000										
# TYPE	RADIUS	DISTANCE	GLASS	INDEX	APE-Y AP	CP	DP	TP	MP (	FLB	
OBJ S	Infinity	0.10000E+21		1.000000	0.00 C	0	0	0	0	0	
1>S	31.9354	4.90200	LAK9	1.694019	17.00* C					0	
2 5	95.0214	0.22600		1.000000	16.36 C					0	
35	18.9471	5.42100	LAK9	1.694019	13.38 C	0	0	0	0	0	
4 S	51.7823	2.82700	SF8	1.694169	12.29 C					0	
5 5	12.8019	6.84900		1.000000	8.58 C	0	0	0	0	0	
STO S	Infinity	6.66300		1.000000	6.17 C	0	0	0	0	0	
7 S	-14.3984	2.00900	F2	1.624088	7.87 C	0	0	0	0	0	
8 5	-257.4193	4.41800	LAK9	1.694019	10.15 C	0	0	0	0	0	
9 S	-20.1304	0.20200		1.000000	10.90 C	0	0	0	0	0	
10 S	149.9510	4.02100	LAK9	1.694019	12.75 C	0	0	0	0	0	
11 S	-42.1828	27.91812		1.000000	13.00* C	0	0	0	0	0	
IMG S	Infinity			1,000000	18.18 C	0	0	0	0	0	
ommand											

Figure 25.2: Select text in the text window. Printing of selected text is performed by clicking on the main menu printer icon (see Fig. 25.3). Note: If no text is selected, the contents of the entire window is printed. See also the CLS command for clearing the text window.

📢 Op T	aliX	-Pro	6.5	5 0:	\op	talix\	exai	nple	s∖Mis	ic\D	OUBLE	_GA	<b>USS-</b> 2	.0
File Li	ist	Edit	Disp	olay	Geor	n.Anal	ysis	Diffr	.Analy	/sis	Tools	Ор	timizati	on
	, 6		3	<b>3</b>	8			<b>N</b>	2 🖓	b	4	7	<b>M</b> #1	IF D
Comma	and :													
			I .											
			Prir	nt w	hol	e tez	xt c	r se	elect	ed	text			

Figure 25.3: Print selected text from the text window. Note: For printing graphics, click on the printer icon at the left bar of each graphics window (see also Fig. 25.4).

#### Send graphics to a file:

```
gra bmp fil c:\graphics.bmp
fan
gra t
```

#### Send graphics with a specified size to a bitmap file:

```
gra bmp fil c:\graphics.bmp
bmpx 1200 ! horizontal with 1200 pixels
bmpy 800 ! vertical height 800 pixels
vie
gra t
```

#### Send text output to printer:

out prn lis out t



Figure 25.4: Print graphics.

### Send text output to printer (short form):

lis > prn

### Send text output to a file:

out fil c:\text.txt
lis
out t

# Macro Language

A macro is a sequence of OpTaliX commands, arithmetic expressions and database item specifications stored in a file. Macro commands may also interactively entered and executed in the command line. There is no functional difference between commands in a command line or stored in a file.

Macros are written to summarize often repeated command sequences into one single command or to enhance the capabilities of OpTaliX with new user-defined or user-specific features.

Creating and executing a macro is a two step process. Macro commands to be used must first be entered in a text file, which has the preferred extension .mac (such as test.mac) but any other extension is also accepted. Editing can be done with any ASCII text editor available under the operating system. OpTaliX offers a built-in macro editor, which avoids the need to invoke an external editor. Up to 20 macros may be edited in the OpTaliX macro editor. The OpTaliX macro editor can be invoked by the command

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or from the menu *Edit* -> *Macro files*.

📢 Macro Editor	_ 🗆 🗙
<u>Eile E</u> dit <u>S</u> earch <u>V</u> iew Run	
<pre>\$pi = %1 rdy s1 = \$pi*sqrt(2) lis print [rdy s1]</pre>	
Macro Parameters: 3.14159	-

Figure 26.1: Macro Editor Window. This example passes one parameter (3.14159) to the macro which is interpreted in the macro script by the %1 token as the first parameter. In the first line of this script, a variable \$pi is defined based on the passed parameter. The second line assigns the value of variable \$pi to the radius of surface 1, multiplied by sqrt(2). The third line list the prescription data and in line 4, radius of surface 1 is output (queried) from the lens database.

After editing the macro sequence, the macro can be immediately executed by clicking on the '**Run**' menu item. External parameters passed to the macro, if required, may be defined in the field labeled

"Macro Parameters:" at the bottom of the macro editor window (see Fig. 26.1). In case a requested %i parameter in the macro script is not available, respectively not defined, it is assumed zero (for numeric values) or blank (for character variables).

The macro editor offers several buffers to hold more than one macro sequence. Selecting the 'File'

-- > 'New' option or by clicking on the icon  $\square$  in the macro editor menu opens a new buffer. Buffers can be selected from the 'View' menu in the macro editor's main menu.

You will be asked at program exit whether to save unsaved buffers or not. Also on closing the macro buffer, either by selecting 'File'  $-i_i$  'Exit' or by clicking on the icon in the upper right corner, a dialog box will request saving of still unsaved macro sequences.

# 26.1 RUN Statement

From the macro editor, the macro can be immediately executed by clicking on the '**Run**' menu in the macro editor window. Alternatively, a saved macro file is executed by the command

```
run filename [parameter1...9]
```

This command reads in and executes the contents of a macro file (given with full path) where [parameter1..9] allows up to 9 expressions (numbers, strings or arithmetic expressions) to be passed to the macro as parameters. Each parameter expression is evaluated and the result (number or string) is substituted for a corresponding special symbol (%1, %2, ... %9) in the macro.

Suppose the following very simple example macro example.mac,

```
! Prints the root of a number
print 'The root of ' %1 'is ' sqrt(%1)
```

which is executed from the command line by

```
run example.mac 2
```

where the number 2 following the macro name is the first parameter to be passed to the macro. The output is

The root of 2.0000000000000 is 1.414213562373095

Note that parameters are not variables, they are essentially constants that are defined at runtime.

# 26.2 Arithmetic Expressions

An expression consists of operands and operators. Operands are constants, lens database items and user defined variables. Operators are

- + addition
- subtraction
- \* multiplication
- / division
- \*\* exponentiation
- ^ exponentiation

There exist also an extensive set of intrinsic functions:

sin(r)	sine of angle in radians
cos(r)	cosine of angle in radians
tan(r)	tangent of angle in radians
exp(x)	$e^x$
log(x)	natural logarithm
log10(x)	common logarithm
logn(n,x)	logarithm base n
sqrt(x)	square root
acos(r)	arccosine
asin(r)	arcsine
atan(r)	arctangent
cosh(r)	hyperbolic cosine
sinh(r)	hyperbolic sine
tanh(r)	hyperbolic tangent
besj0(x)	Bessel function $1^{st}$ kind, order 0
besj1(x)	Bessel function $1^{st}$ kind, order 1
besjn(n,x)	Bessel function $1^{st}$ kind, order n
aint(x)	truncate to a whole number
anint(x)	real representation of the nearest whole number
abs(x)	absolute value
min(a,b)	minimum value
max(a,b)	maximum value
sech(x)	hyperbolic secant ( = $1/cosh(x)$ )
$\operatorname{csch}(x)$	hyperbolic cosecant ( = $1/sinh(x)$ )
rand	random number

Numbers are all assumed to be real and are entered in the usual FORTRAN double precision way. The # sign represents an integer digit.

	Example:
#	1
.#	.1
#.#	1.2
#.#d#	1.2d3
#.#d-#	1.2d-3
#.#d+#	1.2d+3
#.#e#	1.2e3
#.#e-#	1.2e-3
#.#e+#	1.2e+3
#.#D#	1.2D3
#.#D-#	1.2D-3
#.#D+#	1.2D+3
#.#E#	1.2E3
#.#E-#	1.2E-3
#.#E+#	1.2E+3

Note that blank characters are not allowed in arithmetic expressions, except where enclosed in **brackets**. Valid arithmetic expressions are:

print 2+3

```
print (2 + 3)
print ([EFL] + 2)
```

Invalid arithmetic expressions:

print 2 + 3 print [EFL] + 2

# 26.3 Lens Database Items

Macro expressions may include lens database items, which are retrieved from the current optical system. Almost anything that can be entered in the command line has a corresponding lens database item (see also chapter 27 for a complete list of available lens database items). All references to lens database items must be enclosed in rectangular brackets [ and ], even if there are no qualifiers. The syntax for database items mirrors the syntax used for command line input.

For example,

rdy s1 43.5

specifies the curvature on surface 1. The same syntax, but now enclosed in square brackets, without the value 43.5, returns the curvature on surface 1

[rdy s1]

This syntax may be combined with other commands as given in the following examples:

```
thi s2 [EPD] ! sets thickness s2 equal to entrance pupil diameter
cuy s3 -[cuy s4] ! curvature on surface 3 is equal to minus the
! curvature on surface 4
```

Note that the last example (cuy s3 -[cuy s4]) does NOT constitute a permanent functional relationship (or pickup) between the curvatures cuy s3 and cuy s4, it occurs only at the moment of input or macro execution.

Lens database items can be combined with arithmetic operators to form an arithmetic expression anywhere a numeric data entry is expected.

```
fno [EFL]/[EPD] ! sets F-number
thi s3 2*sqrt(3)*[thi s1]
```

As already expressed in section 26.2 above, arithmetic expression must not contain blank characters, except within lens database items or when enclosed in () brackets. For example,

valid: fno [EFL]/[EPD] valid: fno ([EFL] / [EPD]) invalid: fno [EFL] / [EPD]

# 26.4 PRINT Statement

The print statement is used to send data to an output unit (text output window or file). See also section 25 (page 451) for selecting output units and section 26.7 (page 463) for defining formatted output. The print command is followed by a list of expressions. For example,

print 'The entrance pupil diameter is' [epd]

generates the output

The entrance pupil diameter is 12.00000

Strings must be enclosed in quotation marks. Numeric data, being either arithmetic expressions or constants, are output in free floating format displaying full double precision (64 bit) accuracy. The output format can be controlled using the format option as described in section 26.7 (page 463).

Arithmetic expressions are directly solved in print statements. Multiple expressions in an output list may be comma separated. The comma is then repeated in output. For example,

```
$pi = 3.14159
$diam = 10.0
print 'Area of a circle with 10mm diameter = ' $pi*($diam/2)**2 'mm^2'
print 'Some expressions:' 2*[EFL] , atan([NA]), 4*3.14159
```

results in

Area of a circle with 10mm diameter = 78.5397500000000 mm^2 Some expressions: 100.00000000000 , -0.1566953104668687 , 12.5663600000000

Example of changing the output unit in a macro sequence:

out file c:\test.txt	! directs output to file
print 'System focal length' [EFL]	! prints EFL to file
out t	! redirects output to screen (terminal)

If several arithmetic expressions or database items shall be printed in one line, they can be separated by appropriate separators. Valid separators are ',' (comma) or any text enclosed in quotes ' '. Examples:

print 'Two expressions:' [efl], 2\*[bfl]
print 'Two expressions:' [efl] 2\*[bfl]

# 26.5 Formatted Output

The FORMAT statement, when used in conjunction with the print statement, provides explicit information how data and characters are displayed on output. The syntax for defining formatted output closely (but not entirely) follows the conventions of the FORTRAN programming language.

The major difference to the FORTRAN convention is that formatted output is defined by a character string enclosed in apostrophes and appended to the print statement.

Table 26.1: Format Definition				
'format format-items'	Statements for defining the output format must always be enclosed in apostrophes (') or quotes (''). Typically, a format statement is given in conjunction with the print statement. The definition of output formats closely fol- lows the FORTRAN convention. See examples below on how format-items are constructed.			

### Description of format-items:

format-items is a comma-separated list of data-edit-descriptors, (B, O, Z, F, D, E, EN, ES, G, L, A), and control-edit-descriptors (X). The different forms of edit descriptors are described as follows:

Edit Descriptor	Interpretation	Туре
Iw[.m]	Displays value as integer number with field width of w and m	Integer
	digits. Example: I3	
Fw.d	Displays decimal number with field width of $w$ and $d$ decimal	Real
	places, no exponent. Example: The format F8.5 prints the	
	value 12.345 as 12.34500.	
Ew.d	Displays decimal number with field width of w and d deci-	Real
	mal places in exponential representation. Example: The format	
	E12.5 prints the value 12.345 as 0.12345E+02.	
ENw.d	Displays decimal number with field width of w and d deci-	Real
	mal places in engineering notation. Example: The format	
	EN12.5 prints the value 12.345 as 12.34500E+00.	
Gw.d	Displays decimal number in <i>generalized</i> format width of w and	Real or Inte-
	d decimal places. The output format is adapted to optimally	ger
	fit the output width. If necessary, exponential representation is	
	used. Example: The format G12.5 prints the value 0.012345	
	as 0.12345E-01.	
A[w]	Displays alphanumeric field (text string) with a field width of	Character
	w. Example: A10 outputs the string 'This is another exam-	
	ple' as "This is an" without the quotation marks. Longer	
	strings are truncated to width w. Use the "A" format character	
	without the width $(w)$ descriptor if the length of the text output	
	is unknown.	
Zw[.m]	Displays value as hexadecimal number with field width of w	Integer
	and m digits. Example: The format Z4 prints the (decimal)	
	value 43 as 2B in hexadecimal notation.	
Ow[.m]	Displays value as octal number with field width of $w$ and $m$	Integer
	digits.	
nX	Move n spaces right of current position. Inserts space of n	None
	(blank) characters.	

#### Table 26.2: Format Edit Descriptors

#### Example 1:

print 'format F7.3,F10.1' 12.3 14.5

Prints the numeric values (12.3, 14.5) as floating numbers in the formats F7.3 and F10.1. The output is, where \_ represents a blank character (space):

#### Example 2:

```
print 'format F7.3,2X,A12' 12.3 'This is a long text'
prints
```

12.300 This is a lo

because the format descriptor (A12) limits text output to 12 characters. If the length of the output string is not known, use the the generic A format as shown in example 3 below. It will not truncate text output, however, due to the unknown string length, formatted output is not predictable.

#### Example 3:

print 'format F7.3,2X,A,I4' 12.3 'This is a long text' 17

prints

```
12.300 This is a long text 17
```

### 26.6 READ Statement

The READ statement transfers values from an input unit (typically a file) to the variables specified in an input list. Before reading variables from a unit, the input unit must be opened (see OPEN statement) and selected by the SELECT statement. Example:

```
open (unit=1, file='c:\temp\mac_read.txt')
select (1)
read $x $y
close (1)
```

# 26.7 Format Statements defined in Variables

Format definitions may also be stored in variables and re-used for printing data. An example of formatted output is given here:

```
$fmt1 = 'A4,F12.5'
print $fmt1 'formatted number' 4
```

In this example, the format definition is assigned to the variable *\$fmt1*. This variable is then re-used in the print statement in line 2.

# 26.8 CONCATENATION of Strings

The character sequence '//' denotes the concatenation operator. In a command or macro statement, the concatenation operator joins two character strings end to end. For example the strings "sun" and "light" may be concatenated to give "sunlight".

#### **Example 1: Concatenation of Two Strings:**

print 'abc'//'123' outputs the string: 'abc123'

#### **Example 2: Concatenation of String and Variable:**

\$x = 4
print 'abc'//\$x
outputs the string 'abc4'

#### **Example 3: Dynamic File Names:**

do \$x = 1,5
 \$file = 'test'//\$x//'.dat'
enddo

creates the file names

test1.dat test2.dat ... test5.dat

Multiple strings may be concatenated in one line, e.g.

```
print 'abc'//'def'//'ghi'
```

Note that blank strings are considered as "empty" strings according to the OpTaliX syntax definition, i.e. they have no meaning. Accordingly the instruction 'my'//' '//'wife' results in mywife and NOT my wife.

# 26.9 Evaluate Statement "EVA"

The evaluate statement EVA is functionally equivalent to the print statement (see above). It has been included for command compatibility with Code V. In addition to evaluating expressions, the EVA command also supports character strings. For example, the commands

```
print 'The half focal length is' [EFL]/2
eva 'The half focal length is' [EFL]/2
```

are equivalent. The EVA command also evaluates variables and functions such as

eva \$x eva @myfunc

# 26.10 File Inclusion

A file can be included with the command

```
#include filename
```

and the contents of the file "filename" is executed as if it were entered directly in the macro file or on the command prompt. Nesting of included files is permitted to a depth of 10, i.e. an included file itself may call other files via the #include command. For example, consider the macro file "macro1.mac" which calls (includes) the file "macro2.mac"

```
! macrol.mac
#include macro2.mac
print 'Result' pi
```

and

! macro2.mac \$pi = 3.14159

On execution, they are executed as if all macro statements were entered in a single file:

```
! macrol.mac
$pi = 3.14159
print 'Result' pi
```

# 26.11 Variables

Variables are used for temporary storage of values. A variable may contain either a numeric value or a string of characters as data. The length of a variable name can be up to 60 characters. The type of a variable is the type of the data it contains. No distinction is actually made between integer or floating point numbers; all numbers are stored as double precision floating point values. The length of a variable *definition* (arithmetic expression) may be up to 128 characters. String data may also contain up to 128 characters.

Only scalar variables are permitted, that is, only a single value can be stored in a variable. The LVR command (list variables) may be used to display information about the currently defined variables.

LVR	List user-defined variable names and the numeric values associated.
JVR	List user-defined variable names and the numeric values associated.

The default value of an explicitly defined variable is zero (for numeric variables) or an empty string (for string variables).

A variable name **always** begins with a dollar character (\$) followed by at least one alphabetic character, digits or underscores (\_). Spaces are not allowed in variable names. Variable names are case insensitive, that is, \$xy is equivalent to \$XY. The following are examples of valid and invalid variable names.

valid	invalid	
\$x	\$	(at least one alphanumeric character required)
\$xy	\$x y	(space not allowed)
\$a_long_name	х	(missing \$)
\$1a	\$a-b	(arithmetic operators not allowed)

Variables are always declared 'global', that is, a variable is recognized during the entire run of OpTaliX, they can be accessed (set or queried) in all modules (e.g. macros, command line, user-defined graphics, etc) at any time they are required.

Variables may also be combined with qualifiers for surface, field, wavelength or zoom position. For example, a variable definition \$x = 2 may be reused for defining surface, field, wavelengths, zoom positions. With this example \$\$x would define surface \$2. See section 6.2.3, page 36 for more details about this option.

### 26.11.1 Assignment Statement

The assignment statement is used to assign a value to a user-defined variable. The assignment operator (=) must have spaces preceding it and after it. The format of an assignment statement is as follows:

\$user\_var = expression

where

user_var	=	Specifies a user-defined variable name
expression	=	Specifies the value assigned to the variable

#### **Examples:**

\$x = 2	Assigns the value 2.0 to the variable $x$ .
$y = 3 \star x$	Assigns the value $3 \star \$x$ to the variable $\$y$ . The variable $\$x$ must
	have been previously assigned.
\$z = 2*[efl]	Assignment using a lens database item
\$glass = BK7	Assigns the string 'BK7' to the variable \$glass

# 26.12 INPUT Statement

The INPUT statement interrupts the macro execution and prompts the user for numeric data or text data. A dialog box is displayed to enter up to five parameters. Input data is expected from the keyboard only. Up to five variables can be entered simultaneously in a single INPUT statement.

📢 Macro Input F	Macro Input Parameter 🔀					
Enter X and Y	' co	pordinates:				
\$×	:	2				
\$Y	:	3				
Parameter 3	:					
Parameter 4	:					
Parameter 5	:					
Cancel		ОК				

Figure 26.2: Input data

INPUT 'text' \$var1 [\$var2 \$var3 \$var4 \$var5]	Input data in a macro sequence. The command inter- rupts execution of the macro, displays a dialog box for entering the variable(s) and then continues execution of the macro. The parameter 'text' (enclosed in apostro- phes or quotes) is a descriptive text displayed in the dia- log. 'text' is optional and can be omitted. At least one variable (\$var1) must be specified/entered, otherwise the macro will be terminated.
------------------------------------------------------	----------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------------

#### Example 1:

```
input 'Enter x and Y coordinates:' $x $y
print $x $y
```

displays a dialog box for entering the variables \$x, \$y, as shown in Fig. 26.2: Pressing the **OK** button continues execution of the macro, **CANCEL** terminates it.

#### Example 2:

The text field can be omitted, such as

input \$x \$y
print \$x \$y

# 26.13 **OPEN Statement**

The OPEN statement connects an external file to an input/output unit for subsequent read or write. The files are always opened in ASCII format. If a designated file does not exist, it is created.
OPEN (unit = external-file-unit, file = 'filename')	Opens an external file specified by 'filename' and connects it to an input/output unit external file-unit
	The external-file-unit is a scalar INTEGER expression that evaluates to the input/output unit number of an external file. external-file-unit may be any INTEGER number greater than 0. The unit may also be defined in a variable and re-used in the OPEN statement (see example 2 below). filename is a scalar CHARACTER expression, enclosed in apostrophes, that evaluates to the name of a file, including the path specification. Files without path specification are assumed in the directory of the currently loaded optical system. The file name may also be specified in a variable, as shown in example 2 below.
	<pre>Syntax examples: open(unit=3, file='c:\temp\test.txt') open (unit = 1 file = c:\temp\test.txt ) open(unit=\$unit, file=\$file)</pre>
	See also the corresponding statements CLOSE and SELECT.

## Example 1: Writing data to a file:

```
open (unit=1, file='c:\temp\test.txt')
print 'format F10.4,2X,F7.4' EFL BFL
close (1)
```

Example 2: Using variables in OPEN statement:

```
$unit = 4
$file = 'c:\temp\my test file.txt'
open (unit=$unit, file=$file)
print 'some input/output follows'
close ($unit)
```

Note that the unit number 0 (zero) is reserved for the text output window and is not allowed in OPEN and CLOSE statements. See also the SELECT statement for re-directing output to the text output window.

# 26.14 CLOSE Statement

The CLOSE statement terminates the connection between a specified input/output unit number and an external file. The unit must have been opened previously by the OPEN statement.

	Terminates the connection between a specified in- put/output unit number and an external file.
	Examples:
CLOSE (external-file-unit)	close (3) close(\$unit)
	See also the corresponding statements OPEN and SE-LECT.

# 26.15 SELECT Statement

Selects an input/output unit that has been previously opened using the OPEN statement. This statement is particularly useful if more than one unit/file is opened and different operations (read, write) are performed on different files.

SELECT	Selects an input/output unit that has been previously opened using the OPEN statement. Example:
(excernar fife anic)	select (3)

Example 1: Opening more than one unit and selecting the units:

```
open (unit=1, file='input.txt')
open (unit=2, file='output.txt')
select (1)
    print 'Writing text to unit 1'
select (2)
    read $x $y
close (2)
close (1)
```

**Example 2: Selecting units with variables:** 

```
$unit = 1
$screen = 0
open (unit=$unit, file='input.txt')
print $x $y
select ($screen) ! select screen/window (unit 0)
print $x $y   ! print to text window
close ($unit)
```

Note that unit number 0 (zero) is reserved for the text output window. Unit 0 is always opened and need not to be OPENed explicitly. By default, all outputs (PRINT command) are directed to unit 0 (text output window). Only when a output unit other than 0 has been selected and is in use, unit 0 must be explicitly selected in order to write to the text output window. Example:

```
open (unit=37, file='output.txt')
select (37)
```

```
print 'Writing text to unit 37'
select (0)
    print 'other stuff' ! output goes to text output window
close (37)
```

## 26.16 User-defined Functions

A user-defined function is the replacement of a defined name by its corresponding definition. A userdefined function name consists of an at-sign (@) followed by the name. The length of a function name can be up to 60 characters. The function name can have any number of alphabetic characters, digits, and underscores (\_) following the at-sign (@). A special assignment operator (==) must be used for defining functions. The (==) assignment operator cannot have spaces separating the two = signs. A user-defined function assignment (i.e. definition) may include arithmetic expressions and operators (+ - / \* \*\* ^), lens database items or intrinsic functions. The length of a function definition (arithmetic expression) may be up to 128 characters.

### **Examples:**

$\operatorname{Qmy_fkn} == 2 \star [efl]$	! Defines a function name "my_fkn" using a lens database item
$0123 = 12 + \sin(1)$	! Function names may contain digits

### **Invalid Function Definitions:**

@my\_fkn = 2\*[efl] ! Function definition requires two = signs abc == 12+sin(1) ! Function names must start with at-sign (@).

The function definitions may be listed by the LFK command:

LFC	List user-defined function names and the arithmetic definitions associ-
	ated.

Note that the #define form is obsolete and should no longer be used.

## 26.17 Control Statements

Control statements allow the order of execution of statements to be changed. All control statements may be nested.

## 26.17.1 DO Construct

The DO construct specifies the repeated execution (loop) of a block of code. A DO statement begins a DO construct. An ENDDO statement ends the innermost nested DO construct. The maximum nesting depth of DO-ENDDO constructs is 20.

### Syntax:

```
do $user_var = expr1, expr2 [,expr3]
{statements}
```

enddo

#### where:

\$user_var	Specifies a variable reference to contain the loop values.
expr1	Specifies the initial value of the loop variable <pre>\$user_var.</pre>
expr2	Specifies the final value of the loop variable <pre>\$user_var.</pre>
expr3	Optional. Specifies the increment/decrement value of the loop
	variable <pre>\$user_var. If omitted, the default is +1.0. An incre-</pre>
	ment value of 0 is not valid.
{statements}	Specifies the statement(s) to be executed within the DO-ENDDO
	environment.

**Note:** expr1, expr2 and expr3 may contain any valid arithmetic expression using variables, functions or lens database items.

## Example 1:

A simple example indicating the use of arithmetic calculations.

```
do $x = 2,10,2
   $y = 2*$x
   print $x $y
enddo
```

## Example 2:

This example alters the image surface thickness (the defocus) to step through a range of  $\pm 0.1mm$  in increments of 0.02mm. The coupling efficiency (CEF) is printed at the various focal positions.

```
do $x = [thi si]-0.1, [thi si]+0.1, 0.02
    thi s2 = $x
    print $x [cef]
enddo
```

## Example 3:

This example uses macro parameters passed from the command line to the macro. For example the command 'RUN my\_macro.mac 2 10 2' passes the parameter values to be used for %1, %2 and %3 in the following DO-loop:

```
do $x = %1, %2, %3
    print $x
enddo
```

## 26.17.2 WHILE Construct

The WHILE construct specifies the repeated execution (loop) of a block of code until a condition is true. A WHILE statement begins a WHILE construct. An ENDWHILE or ENDDO statement ends the innermost nested WHILE construct. The maximum nesting depth of WHILE-ENDWHILE constructs is 20.

### Syntax:

```
while (while_expr)
   {statements}
```

#### endwhile

In a WHILE loop-control, while-expr is evaluated and if false, the loop terminates. while-expr may contain any valid arithmetic expression using variables, functions or lens database items.

## Example 1:

```
$x = 0
while ($x < 10)
   $x = $x+1
   print $x
endwhile</pre>
```

## Example 2:

```
$x = 0
while ([thi s1] < 5)
   $x = $x+1
   thi s2 $x
   print [mtfa f1]
endwhile</pre>
```

## 26.17.3 IF Construct

The IF construct controls whether a block of statements will be executed based on the value of a logical expression. The syntax of IF constructs is:

```
IF (expr) THEN
{statements}
ELSEIF (expr) THEN
{statements}
ELSE
{statements}
ENDIF
```

where *expr* is a scalar LOGICAL expression. The *statements* are evaluated in the order of their appearance in the construct until a true value is found, or an ELSE statement or ENDIF statement is encountered. If a true value is found, the block immediately following is executed. *Statements* in any remaining ELSEIF statements of the IF construct are not evaluated.

If none of the evaluated expressions is true, then the block of code following the ELSE statement is executed. The ELSE statement and its *statements* must be the last block in the IF construct.

The characters accepted for enclosing IF/ELSEIF expressions are parenthesis () or braces { }.

Logical expressions may include arithmetic expressions (e.g.  $2 \pm \text{sqrt}(\$x)$ ) or database items or a combination of both (such as  $2 \pm [\texttt{efl}]$ ).

IF constructs my be nested. The maximum nesting depth of IF-ELSEIF-ELSE-ENDIF constructs is 20.

## **Rules for constructing Logical Expressions:**

• Logical expressions must be enclosed in () or {} brackets.

- Logical expressions must have a logical operator, such as =, ==, /=, >, >=, <, <=.
- Blank characters are allowed within logical expressions, except within arithmetic expressions. That is,

IF  $(2 \times 2 > 3)$  is correct, whereas

IF ( $2 \times 2 > 3$ ) is not accepted (blanks within arithmetic expression).

### **Operators in IF Expressions:**

The intrinsic operators in IF expressions are:

- = equal to
- == equal to
- /= not equal to
- < less than
- <= less than or equal to
- > greater than
- >= greater than or equal to

## Example 1:

```
$x = 0
if($x > 3) then
    print '$x is greater than 3'
elseif ($x > 0 ) then
    print '$x is greater than 0 but less than 3'
elseif ($x < 0) then
    print '$x is less than zero'
else
    print '$x is zero'
endif</pre>
```

## Example 2:

```
$x = 0
if( [bfl] <= sqrt(100)) then
   $r = 0.5*[rdy s1]
   rdy s3 $r
   print 'Radius at s3 has been adjusted to ' $r
else
   print 'BFL is greater than 10'
endif</pre>
```

## Example 3:

```
if ([gla s2]='n-bk7') then
    print 'true'
else
    print 'false'
endif
```

# 26.18 Return

The return statement passes one or more values from a macro to its caller. A return statement without variables has no effect. Arithmetic expressions are not allowed in the return statement.

## Example 1:

x = sqrt(2)return x ! pass the value of x to the caller

## Example 2:

\$x = sqrt(2)
\$y = sin(1)
return \$x \$y ! pass the values of \$x and \$y to the caller

### Example 3:

```
return ! statement has no effect (variables missing)
return 3*($x+2) ! arithmetic expressions not allwed in return statement!
```

## 26.19 Comments

The character ! indicates a comment except where it occurs in a character context. Examples:

```
a = 3 ! this is a comment, which is not processed print 'variable a ' a ! this prints the variable
```

# 26.20 Logical Line Separation

The character ; separates logical lines on a single physical line. For example,

```
THI s1..3 12 ; LIS; fan
```

is processed as if the following lines were entered separately

```
THI s1..3 12
LIS
fan
```

# 26.21 Logical Line Continuation

The character & as the last non-blank character of a line signifies that the logical line is continued on the next physical line. <sup>1</sup> If a character context in a macro file is being continued, the & may not be followed by a comment. If the first non-blank character is &, then the continuation begins at the character position immediately following the &; otherwise it begins in column 1.

### **Example:**

```
The first line will be & continued by a second line
```

<sup>&</sup>lt;sup>1</sup>Note that the & character continues lines *only* in macro files. It has a different meaning in the command line, where it invokes option dialog boxes for commands.

## is interpreted as a single line:

The first line will be continued by a second line

# 27

# **Lens Database Reference**

This chapter summarizes the available lens database items. Almost all commands have a corresponding lens database item. The syntax for lens database items is identical to the syntax used in the command line. Unless otherwise noted, the returned quantity is a numeric value.

When specifying lens database items, the same mnemonics and syntax is used in the command line, in a macro file or as constraint/target in the definition of the optimization merit function. Lens database items must always enclosed in square brackets, [ and ]. Examples of valid and invalid lens database items are

[thi s3]	valid					
thi s3	invalid,	brackets	missi	ng		
[EFL]	valid					
[EFL ]	valid					
[E F L ]	invalid,	keywords	must	not	include	blanks

Lens database items can also be used in arithmetic expressions such as

```
thi s3 sqrt(2*[SYL]+3.14159)
```

Lens database items can be printed via the print command. For example,

```
print 'Radius = ' [rdy s3]
```

outputs the radius of curvature on surface 3.

Lens database items accept variables in conjunction with qualifiers (for surface, field, wavelength, zoom, etc), such as

thi s\$var 10.5

where var is the integer value of variable var. Assuming var = 3, this syntax may be understood as concatenating "s" (without the quotes) and the integer value of var to form the string "s3".

Configuration Data:		
REF [zk]	Reference wavelength number	
WL wk [zk]	Wavelength at wavelength number wk, zoom position zk	
	continued on next page	

continued from previous page			
NWL	Number of wavelength defined in the system		
XAN fi [zk]	X-angle (in degree) for field number fi and (optional) zoom po-		
	sition zk. Note: If XAN is not the field specification value, for		
	example when XIM defines the X-field, XAN returns the paraxial		
	equivalent to the field specification. XAN = $tan^{-1}$ (XIM/EFL).		
YAN fi [zk]	Y-angle (in degree) for field number fi and (optional) zoom po-		
	sition zk. See also the note given for XAN		
YOB fi [7k]	$X_{\text{object height for field number finand (optional) zoom position}$		
	$x$ -object height for heid handler $\pm \pm$ and (optional) zoom position		
VOR fi [ak]	V object height for field number fi and (optional) zoom position		
IOB II [ZK]	1-object height for heid humber 11 and (optional) zoom position		
XTM 64 [-]-]	ZR. See also the note given for AAN.		
XIM II [ZK]	A-Image neight (paraxia) for neid number 11 and (optional)		
	zoom position $z_{k}$ . See also the note given for XAN.		
YIM İl [zk]	Y-image height (paraxial) for field number f1 and (optional)		
	zoom position zk. See also the note given for XAN.		
NFI	Number of fields defined in the system		
FNO [zk]	Paraxial F-number		
NA [zk]	Numerical aperture in image space		
NAO [zk]	Numerical aperture in object space		
EPD [zk]	Entrance pupil diameter		
APD [zk]	Exit pupil diameter <sup>1</sup>		
PUI	Intensity apodization across pupil		
PUX	Apodization relative X-pupil coordinate at which PUI is reached		
PUY	Apodization relative Y-pupil coordinate at which PUI is reached		
	Paraxial Data:		
EFL [zk]	Equivalent focal length, Y/Z-cross section, default		
EFLX [zk]	Equivalent focal length, X/Z-cross section		
DEFL [zk]	Differential EFL (based on differential rays), only at infinity ob-		
	ject distance.		
PWR [zk]	Optical power = $1/EFL$		
MFL sk	Module focal length		
BFL [wk] [zk]	Back focal length, if wk is absent, reference colour is used.		
OAL [sij] [zk]	Overall length between surface vertices si to si		
SYL [sii] [zk]	Overall length between surface vertices si to si. Without surface		
	qualifier first surface to image plane is returned		
SH1 [zk]	Position of front principal plane measured from vertex of first sur-		
	face		
SHO [7k]	Position of rear principal plane measured from vertex of last sur-		
	face		
	1400.		
	Overall length ( - object image distance for finite conjugates, re-		
OAL [zk]	Overall length (= object-image distance for finite conjugates, re-		
OAL [zk]	Overall length ( = object-image distance for finite conjugates, re- spectively first surface to image for infinite object distance)		
OAL [zk] OID [zk]	Overall length ( = object-image distance for finite conjugates, re- spectively first surface to image for infinite object distance) Object to image distance		
OAL [zk] OID [zk] MAG [zk]	Overall length ( = object-image distance for finite conjugates, re- spectively first surface to image for infinite object distance) Object to image distance Magnification		

<sup>1</sup>APD is derived from the German word 'Austrittspupillendurchmesser' = exit pupil diameter.

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Differential magnification (based on differential rays)
Reduction factor (= -MAG)
Entrance pupil diameter
Location of exit pupil from last surface
1/SAP
Location of entrance pupil from first surface
Pupil relay distance (distance of entrance pupil to exit pupil)
1/PRD
Paraxial direction angle of the marginal aperture ray
same as UMY
Paraxial height of the marginal aperture ray
same as HMY
Paraxial direction angle of chief ray
same as UCY
Paraxial height of chief ray
same as HCY
Surface Data:
Number of object surface, returns an integer value. Example: eva
[so]
Number of stop surface, returns an integer value. Example: eva
[ss]
Number of image surface, returns an integer value. Example: eva
[si]
Thickness on surface sk, zoom position zk
Reference thickness on surface sk
Image distance (THI si-1) at zoom position zk
Image clearance, the smaller distance (edge or axis) between sur-
face $i-1$ and the image surface $i$ .
Index of refraction at surface sk, wavelength wk.

UMY sk [zk]	Paraxial direction angle of the marginal aperture ray
UA sk [zk]	same as UMY
HMY sk [zk]	Paraxial height of the marginal aperture ray
HA sk [zk]	same as HMY
UCY sk [zk]	Paraxial direction angle of chief ray
UB sk [zk]	same as UCY
HCY sk [zk]	Paraxial height of chief ray
HB sk [zk]	same as HCY
	Surface Data:
SO	Number of object surface, returns an integer value. Example: eva
	[so]
SS	Number of stop surface, returns an integer value. Example: eva
	[ss]
si	Number of image surface, returns an integer value. Example: eva
	[si]
THI sk [zk]	Thickness on surface sk, zoom position zk
THR sk [zk]	Reference thickness on surface sk
IMD [zk]	Image distance (THI si-1) at zoom position zk
IMC [zk]	Image clearance, the smaller distance (edge or axis) between sur-
	face i-1 and the image surface i.
IND sk wk	Index of refraction at surface sk, wavelength wk.
CUX sk [zk]	Curvature in X/Z plane
CUY sk [zk]	Curvature in Y/Z plane
RDX sk [zk]	Radius of curvature in X/Z plane
RDY sk [zk]	Radius of curvature in Y/Z plane
, , , , ,	
ADE SK [ZK]	Tilt angle (in degree) around X-axis
BDE SK [ZK]	Tilt angle (in degree) around Y-axis
CDE SK [ZK]	Tilt angle (in degree) around Z-axis
XDE SK [ZK]	X-decenter
YDE SK [ZK]	Y-decenter
ZDE SK [ZK]	Z-decenter
AADE sk [zk]	Tilt angle (in degree) of array cells around local X-axis
ABDE sk [zk]	Tilt angle (in degree) of array cells around local Y-axis
ACDE sk [zk]	Tilt angle (in degree) of array cells around local Z-axis
[]	
XSG sk [zk]	Global vertex X-coordinate of surface sk. Coordinates are al-
	ways referred to the global system.
	continued on next page

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DMAG [zk]

RED [zk]

EPD [zk]

SAP [zk] SAPI [zk]

SEP [zk]

PRD [zk]

PRDI [zk]

continued from previous page				
YSG sk [zk]	Global vertex Y-coordinate of surface sk. Coordinates are always			
	referred to the global system.			
ZSG sk [zk]	Global vertex Z-coordinate of surface sk. Coordinates are always			
	referred to the global system.			
XSC sk [zk]	Global vertex X-coordinate of surface sk. Coordinates are re-			
	ferred to the coordinate system defined by the GLO sk command			
	Compare with XSG command above			
VSC ob [zk]	Clobal wartax V coordinate of surface ale Coordinates are re-			
ISC SK [ZK]	formed to the appording to sustain defined by the CLO sk command			
	Compare with VSC command shouse			
	Children and So command above.			
ZSC SK [ZK]	Global vertex Z-coordinate of surface sk. Coordinates are re-			
	ferred to the coordinate system defined by the GLO sk command.			
	Compare with ZSG command above.			
CXG sk [zk]	global X-direction cosine of surface normal			
CYG sk [zk]	global Y-direction cosine of surface normal			
CZG sk [zk]	global Z-direction cosine of surface normal			
	Ath order aspheric constant			
A SK [ZK]	4 h order aspheric constant			
D SK $[2K]$	$S^{t}h$ order aspheric constant			
	$\delta^{*}n$ order aspheric constant			
D SK [ZK]	$10^{t} n$ order aspheric constant $12^{t} h$ order aspheric constant			
E SK [ZK]	$12 n$ order aspheric constant $14^{th}$ order aspheric constant			
F SK [ZK]	14 <i>n</i> order aspheric constant $16^{t}$ h order aspheric constant			
G SK [ZK]	$10^{th}$ order aspheric constant			
H SK [ZK]	Conie constant			
K SK [ZK]	Come constant			
SAG sk x_height	Surface sag at surface sk. x_height and y_height are the			
y_height	local coordinates at the tangent plane of surface sk.			
DEF	Defocus			
	Arrays:			
ARX sk	Array surface X-spacing			
ARY sk	Array surface Y-spacing			
ARXO sk	Array surface X-offset of entity of array channels			
ARYO sk	Array surface Y-offset of entity of array channels			
AMX sk	$\pm$ limit for grid in X-direction			
AMY sk	$\pm$ limit for grid in Y-direction			
AADE sk	$\alpha$ -tilt angle (in degree) of each array cell.			
ABDE sk	$\beta$ -tilt angle (in degree) of each array cell.			
ACDE SK	$\gamma$ -tilt angle (in degree) of each array cell.			
	Grating/Hologram:			
GRU SK	Grating order			
GRA SK	Grating frequency X (grooves per mm)			
GKI SK	Grating frequency r (grooves per mm)			
HWL SK	noiogram design wavelength (in $\mu m$ )			
	continued on next page			

r

continued from previous page		
Materials Data:		
GLA sk [zk]	Returns string with glass name	
GL1 sk [zk]	Returns string with glass name, equivalent to GLA	
GL2 sk [zk]	Returns string with glass name on "right" side of surface	
EXC sk [zk]	Linear expansion coefficient $\cdot 10^6$	
DNO sk [zk]	Offset on refractive index	
DVO sk [zk]	Offset on Abbe number (V-number)	
GADE sk [zk]	Tilt of GRIN profile around X-axis	
GBDE sk [zk]	Tilt of GRIN profile around Y-axis	
GCDE sk [zk]	Tilt of GRIN profile around Z-axis	
GXDE sk [zk]	X-decenter of GRIN profile	
GYDE sk [zk]	Y-decenter of GRIN profile	
	1	
ABBE sk	Abbe number at surface sk.	
DNDT sk wk [TEMP PRE]	Absolute dndT at surface sk, wavelength wk. The absolute dndT	
- L J	is referred to vacuum (the default in $OpTaliX$ if temperature cal-	
	culations are concerned). Optional parameters are Temperature	
	TEMP (in °C) and pressure PRE (in mmHg). If not specified.	
	TEMP defaults to 20°C and PRE to 760 mmHg.	
ADNDT sk wk [TEMP	Absolute dndT at surface sk, wavelength wk. The absolute dndT	
PREI	is referred to vacuum. ADNDT is a complementary command to	
]	DNDT (see above).	
RDNDT sk wk [TEMP	Relative dndT at surface sk, wavelength wk, RDNDT is referred	
PREI	to air. See also the relation between absolute dndT and relative	
-	dndT in section 13.2, page 223.	
EXC sk	Linear expansion coefficient. Unit = $*10^6$ . at surface sk.	
EXM sk	Linear expansion coefficient of mirror substrate at surface sk.	
	Unit = $*10^{6}$ .	
SPG sk	Specific gravity $[g/cm^2]$ at surface sk.	
RHO sk	Specific gravity, alternative command to SPG, at surface sk.	
Apertures:		
CIR sk pk [zk]	Circular aperture radius of surface sk, pupil number pk, zoom	
	position zk	
REX sk pk [zk]	Rectangular aperture, X-extension	
REY sk pk [zk]	Rectangular aperture, Y-extension	
ELX sk pk [zk]	Elliptical aperture, half X-axis	
ELY sk pk [zk]	Elliptical aperture, half Y-axis	
ADX sk pk [zk]	Aperture decenter X, $pk = pupil number$	
ADY sk pk [zk]	Aperture decenter Y, $pk = pupil number$	
ARO sk pk [zk]	Aperture rotation (in degree)	
SD sk [fij] [zij]	Maximum semi-diameter on surface sk. In absence of field and	
	zoom qualifiers, value is calculated at all fields and zoom posi-	
	tions.	
WTA [zk]	Weight on aperture (used in optimization only)	
	Environmental Data:	
TEM sk [zk]	Temperature (in $^{\circ}C$ )	
	continued on next page	

continued from previous page		
PRE sk [zk]	Pressure (in mm Hg)	
	Ray Data:	
AOI sk fi zi wi [zk] rel_apeX rel_apeY	Angle of incidence of a ray at surface si, field fi, zoom position zi, wavelength wi. The values rel_apeX, rel_apeY are the relative coordinates in the entrance pupil. The result is in degree. Note that all parameters are obligatory. Example: aoi s3 f5 w1 0 1 < 15	
AOR sk fi zi wi [zk] rel_apeX rel_apeY	Angle of refraction (or reflection) of a ray with respect to the local surface normal. All parameters, surface sk, field fi, zoom position zi, wavelength wi are obligatory. The values rel_apeX, rel_apeY are the relative coordinates in the entrance pupil. The result is in degree. Example: aor s3 f5 w1 0 1 < 15.	
AOE sk fi zi wi [zk] rel_apeX rel_apeY	Angle of exit of a ray with respect to the local surface normal. Note that this command is synonymous the the AOR command given above. All parameters, surface sk, field fi, zoom posi- tion zi, wavelength wi are obligatory. The values rel_apeX, rel_apeY are the relative coordinates in the entrance pupil. The result is in degree. Example: aoe s3 f5 w1 0 1 < 15.	
X sk wk fk rx ry [zk] [gk] Y sk wk fk rx ry [zk] [gk]	X-intersection coordinate of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry Y-intersection coordinate of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry	
Z sk wk fk rx ry [zk] [gk]	Z-intersection coordinate of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry	
XGR wij fk [zk] YGR wij fk [zk]	X-coordinate of spot gravity center on the image surface for wave- length range wij, field fk Y-coordinate of spot gravity center on the image surface for wave- length range wij, field fk	
CX sk wk fk rx ry [zk] [gk] CY sk wk fk rx ry [zk] [gk] CZ sk wk fk rx ry [zk] [gk] CXG sk wk fk rx ry [zk] CYG sk wk fk rx ry [zk] CZG sk wk fk rx ry [zk]	X-direction cosine of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry Y-direction cosine of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry Z-direction cosine of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry Global X-direction cosine of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry Global Y-direction cosine of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry Global Z-direction cosine of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry Global Z-direction cosine of ray on surface sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry	
CXN sk wk fk rx ry [zk]	X-direction cosine of surface normal on intersection of ray at sur- face sk, wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry continued on next page	

continued from previous page		
CYN sk wk fk rx ry	Y-direction cosine of surface normal on intersection of ray at sur-	
[zk]	face sk, wavelength wk, field fk, relative x-pupil rx, relative	
	y-pupil ry	
CZN sk wk fk rx ry	Z-direction cosine of surface normal on intersection of ray at sur-	
[zk]	face sk, wavelength wk, field fk, relative x-pupil rx, relative	
	y-pupil ry	
NRAYS wk fk [zk]	Number of rays traced at wavelength wk, field fk, and optional	
	zoom position zk.	
	Polarization Data:	
POLX fk wk sk rel_apeX	Polarization amplitude component X for a single ray at field fk,	
rel_apeY	wavelength wk, surface sk.	
POLY fk wk sk rel_apeX	Polarization amplitude component Y for a single ray at field fk,	
rel_apeY	wavelength wk, surface sk.	
POLP fk wk sk rel_apeX	Polarization phase (difference) for a single ray at field fk, wave-	
rel_apeY	length wk, surface sk. The polarization phase is given in radians.	
POLD fk wk sk rel_apeX	Degree of polarization for a single ray at field $fk$ , wavelength $wk$ ,	
rel_apeY	surface sk.	
	Tolerance/Sensitivity Data:	
TSF [fk fij	Tolerance sensitivity on test-plate fit. Assumes that a tolerance	
wk wij] sk sij	has been defined on the corresponding surface in the tolerance	
	editor. See the command DLF or a description of test plate fit on	
	page 411. If a tolerance on this parameter has not been defined in	
	the tolerance editor, the program assumes DLF 2.0 (fringes) for	
	calculating tolerance sensitivity TSF.	
TSI [fk fij	Tolerance sensitivity on surface irregularity. Assumes that a tol-	
wk wij] sk sij	erance has been defined on the corresponding surface in the toler-	
	ance editor. See the command IRR on page 407. If a tolerance on	
	this parameter has not been defined in the tolerance editor, the pro-	
	gram assumes IRR 0.4 (fringes) for calculating tolerance sensi-	
	tivity TSI.	
TST [fk fij	Tolerance sensitivity on surface thickness (distance). Requires	
wk wij] sk sij	that a tolerance has been defined on the corresponding surface	
	in the tolerance editor. See the command DLT on page 407. If a	
	tolerance on this parameter has not been defined in the tolerance	
	editor, the program assumes DLT 0.02 for calculating tolerance	
	sensitivity TST.	
TSN [fk fij	Tolerance sensitivity on index of refraction. Requires that a toler-	
wk wij] sk sij	ance has been defined on the corresponding surface in the toler-	
	ance editor. See the command DLN, page 407, for defining index	
	tolerances. If a tolerance on this parameter has not been defined	
	in the tolerance editor, the program assumes DLN 0.001 for cal-	
	culating tolerance sensitivity TSN.	
	continued on next name	
	continued on next page	

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TSV [fk fij wk wij] sk sij	Tolerance sensitivity on dispersion. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLN, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLV 0.008 (0.8%) for calculating tolerance sensitivity TSV.
TSX [fk fij wk wij] sk sij	Tolerance sensitivity on X-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLX, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLX 0.02 (mm) for calculating tolerance sensitivity TSX.
TSY [fk fij wk wij] sk sij	Tolerance sensitivity on Y-decenter. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLY, page 407, for defining dispersion toler- ances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLY 0.02 (mm) for calculating tolerance sensitivity TSY.
TSZ [fk fij wk wij] sk sij	Tolerance sensitivity on Z-decenter. A Z-decenter is equivalent to a thickness tolerance. Requires that a tolerance has been de- fined on the corresponding surface in the tolerance editor. See the command DLZ, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLZ 0.05 (mm) for calculating tol- erance sensitivity TSZ.
TSA [fk fij wk wij] sk sij	Tolerance sensitivity on tilt about X-axis. Requires that a toler- ance has been defined on the corresponding surface in the toler- ance editor. See the command DLA, page 407, for defining dis- persion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLA 5 (ar- cmin) for calculating tolerance sensitivity TSA.
TSB [fk fij wk wij] sk sij	Tolerance sensitivity on tilt about Y-axis. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLB, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLB 5 (arcmin) for calculating tolerance sensitivity TSB.
TSG [fk fij wk wij] sk sij	Tolerance sensitivity on tilt about Z-axis. Requires that a tolerance has been defined on the corresponding surface in the tolerance editor. See the command DLG, page 407, for defining dispersion tolerances. If a tolerance on this parameter has not been defined in the tolerance editor, the program assumes DLG 5 (arcmin) for calculating tolerance sensitivity TSG.
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TSH [fk fij	Tolerance sensitivity on index homogeneity. Requires that a tol-	
wk wij] sk sij	erance has been defined on the corresponding surface in the tol-	
	erance editor. See the command HOM, page 407, for defining	
	homogeneity tolerances. If a tolerance on this parameter has not	
	been defined in the tolerance editor, the program assumes HOM	
	50 $(50 \cdot 10^{-6})$ for calculating tolerance sensitivity TSH.	
	Geometric Analyses:	
SPD fk wk [zk]	Spot diameter (rms)	
SPX fk wk [zk]	Spot diameter (rms), only X-direction	
SPY fk wk [zk]	Spot diameter (rms), only Y-direction	
SPDPV fk wk [zk]	Spot diameter (PV)	
SPXPV fk wk [zk]	Spot diameter (PV), in X-direction	
SPYPV fk wk [zk]	Spot diameter (PV), in Y-direction	
LAC fk [wij] [zk]	Lateral colour	
LAX fk wk [zk]	Logitudinal aberration X	
ape_relX ape_relY		
LAY fk wk [zk]	Logitudinal aberration Y	
ape_relX ape_relY		
SSR [wij] [zij]	Secondary spectrum, weighted rms-value.	
SPA [zk]	$3^{rd}$ order spherical aberration	
COMA [zk]	$3^{rd}$ order coma	
ASTI [zk]	$3^{rd}$ order astigmatism	
PETZ [zk]	$3^{ra}$ order petzval sum (field curvature)	
PTZ [zk]	synonymous to PETZ, $3^{rd}$ order petzval sum (field curvature), for	
	Code V compatibility only.	
DIST [zk]	$3^{ra}$ order distortion	
DST [zk]	synonymous to DIST, $3^{ra}$ order distortion, for Code V compati-	
	bility only.	
LCA [zk]	3 <sup><i>ra</i></sup> order longitudinal colour	
TCA [zk]	$3^{ra}$ order transversal colour	
AX [zk]	synonymous to TCA, $3^{ra}$ order longitudinal colour, for Code V	
	compatibility only.	
DISX İK [ZK]	Distortion, X-direction	
DISY ik [zk]	Distortion, Y-direction	
FDISX fk [zk]	F-theta distortion, X-direction	
FDISY IK [ZK]	F-theta distortion, Y-direction	
VIG [İK] [ZK]	Vignetting factor relative to field 1. Values are returned between	
	U (100% vignetting) and 1 (no vignetting).	
ECG IK [W1]] dlam_x	Encircled energy (geometric) contained in image area $X =$	
	$alam_x, Y = alam_y$	
GMTET [IK ZK]	Tangenual geometric MTF at field fk, zoom position zk.	
GMIES [IK ZK]	Sagiual geometric Wilf at field IK, zoom position ZK.	
GMIFA [IK ZK]	Average geometric MTFA = $0.5 \text{ (CMTFT} + \text{CMTFC})$	
	U.5 (GMTET + GMTES)	
	continued on next page	

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ASTT fk wk rx ry [zk]	Tangential astigmatism along a single ray defined by wavelength wk, field fk, relative x-pupil rx, relative y-pupil ry. Astigma-		
	tism is always measured at the image surface. If wk is omitted,		
	the RMS value over all wavelengths is returned.		
ASTS fk wk rx ry [zk]	Sagittal astigmatism along a single ray defined by wavelength wk,		
	field fk, relative x-pupil rx, relative y-pupil ry. Astigmatism is		
	always measured at the image surface. If wk is omitted, the RMS		
	value over all wavelengths is returned.		
ASTD fk wk rx ry [zk]	Astigmatic difference along a single ray defined by wavelength		
	wk, field fk, relative x-pupil rx, relative y-pupil ry. Astigma-		
	tism is always measured at the image surface. If wk is omitted,		
	The RIVIS value over all wavelengths is returned.		
	Iransmission Analyses:		
TRA İK WK SK ZK	Mean (average) transmission along a single ray, defined at field fk,		
pupil_X, pupil_Y	wavelength number wk, zoom position zk. The data pair (pupil_x,		
	$pupil_Y$ defines the relative coordinates in the entrance aperture.		
IRAS IK WK SK ZK	S-poi transmission along a single ray, defined at field ik, wave-		
pupii_x, pupii_i	rength humber wk, zoom position zk. The data pair (pupil_x,		
	<b>D</b> pupil <b>i</b> ) defines the relative coordinates in the entrance aperture.		
IRAP IK WK SK ZK	length number wk zoom position zk. The date pair (pupil x		
pupii_x, pupii_i	pupil V) defines the relative coordinates in the entrance enerture		
	Diffraction A polyses:		
	Fiber coupling officiency		
CEF [IK WK ZK]	Fiber coupling efficiency in decibel		
CEPDE [IK WK ZK]	Strehl ratio		
DMD [fk fi i	Conrady D-d sum at field fk weighted over wavelengths wiji		
wklwi, il ape x ape v	See also sect 14.2.12		
MTF fk [wii] [zk]	Mean MTF = $0.5*$ MTF(Sag+Tan). Equivalent to the MTFA com-		
	mand (see below).		
MTFA fk [wii] [zk]	Average (mean) MTF = $0.5*$ MTF(Sag+Tan)		
MTFS fk [wij] [zk]	Sagittal MTF		
MTFT fk [wij] [zk]	Tangential MTF		
WAV fk wk [zk]	Wavefront aberration (rms)		
WAVPV fk wk [zk]	Wavefront aberration, peak-to-valley (PV)		
WAVZ fk wk [zk]	Wavefront aberration (rms), with selected Zernike terms sub-		
	tracted. Define Zernike terms by the ZWACT command, see page		
	150.		
PSDX fk [zk]	PSF width-x at intensity-threshold at field fk.		
[threshold]			
PSDY fk [zk]	PSF width-y at intensity-threshold at field fk.		
[threshold]			
PSE fk [zk]	Ellipticity of PSF, ratio of PSDX/PSDY at intensity-threshold		
[threshold]	at field fk.		
ECE fk diam	encircled energy within diameter (diam) at field fk.		
EQE fk diam	ensquared energy within diameter (diam) at field fk.		
KEFS fk	Knife Edge Function (KEF) in the sagittal orientation at field fk.		
	continued on next page		

continued from previous page		
KEFT fk	Knife Edge Function (KEF) in the tangential orientation at field	
	fk.	
	Gaussian Beams:	
WRX [sk]	Gaussian beam waist radius X (in mm) at surface sk	
WRY [sk]	Gaussian beam waist radius Y (in mm) at surface sk	
ZWX [sk]	Location of Gaussian beam waist X relative to surface sk	
ZWY [sk]	Location of Gaussian beam waist Y relative to surface sk	
RCX [sk]	Radius of X-curvature of Gaussian beam waist at surface sk	
RCY [sk]	Radius of Y-curvature of Gaussian beam waist at surface sk	
SRX [sk]	Spot size of Gaussian beam in X/Z-plane at surface sk	
SRY [sk]	Spot size of Gaussian beam in Y/Z-plane at surface sk	
GDX [sk]	Divergence of Gaussian beam in X/Z-plane at surface sk. Must	
	have the Gaussian source parameters WRX, WRY, RCX, RCY	
	properly set.	
GDY [sk]	Divergence of Gaussian beam in Y/Z-plane at surface sk. Must	
	have the Gaussian source parameters WRX, WRY, RCX, RCY	
	properly set.	
RRX [sk]	Rayleigh range of Gaussian beam in X/Z-plane at surface sk.	
RRY [sk]	Rayleigh range of Gaussian beam in Y/Z-plane at surface sk.	
	Fiber Data:	
FSR [zk]	Source fiber mode field radius (in mm)	
FSD [zk]	Source fiber far-field divergence (in rad)	
FSA [zk]	Fiber source $\alpha$ -tilt in degree	
FSB [zk]	Fiber source $\beta$ -tilt in degree	
FSN1 [zk]	Source fiber, index of refraction $n_1$ of core material	
FSN2 [zk]	Source fiber, index of refraction $n_2$ of cladding material	
FSCR [zk]	Source fiber, core radius in mm	
FRR [zk]	Receiving fiber mode field radius (in mm)	
FRD [zk]	Receiving fiber far-field divergence (in rad)	
FRA [zk]	Receiving fiber $\alpha$ -tilt in degree	
FRB [zk]	Receiving fiber $\beta$ -tilt in degree	
FRX [zk]	Receiving fiber x-offset (in mm) with respect to the chief ray	
FRY [zk]	Receiving fiber y-offset (in mm) with respect to the chief ray	
FRN1 [zk]	Receiving fiber, index of refraction $n_1$ of core material	
FRN2 [zk]	Receiving fiber, index of refraction $n_2$ of cladding material	
FRCR [zk]	Receiving fiber, core radius in mm	
Illumination Source Data:		
SUSE sk 0 1	Use illumination source k (0=no, 1=yes). Example, enabling	
	source 2: suse s2 1	
SPWR sk pwr	Source power	
SXEX sk x_extension	Source X-extension (full width)	
SYEX sk y_extension	Source Y-extension (full width)	
SXDE sk x_dec	Source X-decenter	
SYDE sk y_dec	Source Y-decenter	
SZDE sk z_dec	Source Z-decenter	
SADE sk alpha	Source tilt ( $\alpha$ ) about X-axis	
SBDE sk beta	Source tilt ( $\beta$ ) about Y-axis	
	continued on next page	

continued from previous page	
SCDE sk gamma	Source tilt ( $\gamma$ ) about Z-axis
SARAY sk analysis_rays	Source: Number of analysis rays
SPRAY sk plot_rays	Source: Number of plot rays
SGREF sk O G	Source reference: $O = object$ , $G = global$
SDIVX sk x_div	Source divergence X (in degrees), full width
SDIVY sk y_div	Source divergence Y (in degrees), full width
SOFA sk x_offs	Source emittance angular offset in Y direction (in degrees)
SOFB sk y_offs	Source emittance angular offset in X direction (in degrees)
	Illumination Analysis Data:
RPWR	Return received power, including all activated sources
EPWR	Return emitted power, all activated sources
NILR	Return number of successfully received rays at target surface, in-
	cluding all active sources.
	Miscellaneous Functions
RAIS	Ray aiming maximum step relative to entrance pupil (default = 1).
RAIT	Ray aiming tolerance relative to entrance pupil (default = $0.001$ ).
	Returns 80 character string containing lens title.
COM sk	Returns the comment string for surface sk
	Returns 12-character string with current date in the format DD
	MMMM .T.T.T.T
ТТМ	Returns 8-character string with current time in the format
FNAME	Returns a character string containing the file name (without nath)
FDNAME	Returns a character string containing the file path + name
FDATH	Returns a character string containing the file path only
POX [7k]	Plot offset X in paper units
	Plot offset V in paper units
	Plot offset 7 in paper units
	Weight (in grams)
SPC [ak]	Specific gravity (in $a/cm^3$ )
DIANCK WANAL T	Specific gravity (in $g/ch^2$ ) Calculate radiance of a black body source according to Planck's
I LANCK WAVEL I	law ways of a black body source according to Hanck's
	Taw. Waver is the wavelength in $\mu m$ , i is the temperature in Kalvin
	Kelvili.
INDY [fle set dlam]	Lateral dispersion in V direction given at the image surface
LADA [IK WK GIAM]	Draferably used in spectrometric systems. Calculates the spread
	of a wavelength interval dlam (in um) at the image surface
	of a wavelength interval dram (in $\mu m$ ) at the image surface.
	Example. 140x 11 w2 0.01 calculates the spatial extension (approad) of the wavelength interval $A$ ) = 0.01 was in the image
	(spread) of the wavelength interval $\Delta \lambda = 0.01 \mu m$ in the image.
	The resulting unit is $\mu m/m n$ .
LADY [IK WK dlam]	Lateral dispersion in Y-direction, given at the image surface.
	of a wavelength integral allow (in www) at the inverse of
	of a wavelength interval $\alpha_{\perp}$ am (in $\mu m$ ) at the image surface.
	Example: $1 \text{ ady } 11 \text{ w} 2 \text{ 0.01}$ calculates the spatial extension
	(spread) of the wavelength interval $\Delta \lambda = 0.01 \mu m$ in the image.
	The resulting unit is $\mu m/mm$ .
[ RAND [SEED num]	Random number. Optionally the seed can be set by "RAND SEED
	num", where num is any arbitrary number.

# **Colour Names**

28

This chapter describes names of predefined colours in OpTaliX to be used in most graphical output. Currently colours can be separately defined for fields, coatings and encircled energy geometric (ECG). In later versions this will also be possible for wavelengths and zoom positions.

Colours for various plot/analysis types are specified by the CLS command. For a detailed description see the individual sections on page 47 (fields), page 390 (coatings).

Note that colour settings are preserved for a specific optical design. On loading (restoring) a new design, colours are set to their default values unless user-defined colours are specified in the new file.

## **28.1** Predefined colours

Predefined colours are designated by names. The first three characters are significant in specifying colour names.

Short name	colour	RGB - value
RED	red	255,0,0
GRE	green	0,255,0
BLU	blue	0,0,255
MAG	magenta	255,0,255
CYA	cyan	0,255,255
YEL	yellow	255,255,0
BLA	black	0,0,0
BRO	brown	185,92,0
ORA	orange	255,128,0
GRY	grey	192,192,192
VIO	violet	192,128,255
TUR	turquoise	0,194,194
SAL	salmon	255,128,128

# **28.2 Default Colours in Field Plots**

The default sequence of colours for field is RED, GREEN, BLUE, MAGENTA, and CYAN. This sequence is repeated up to the last field for systems with more than 5 fields. Use the CLS FLD command (see page 47) to specify your own field colours.

# **28.3** Default Colours in Coating Analysis

Default colours used in coating analysis plots are RED GREEN BLUE.Use the CLS COA command (see page 390) to specify your own colours.

# 28.4 Default Colours in Encircled Energy Geometric (ECG) Analysis

Default colours used in encircled energy geometric (ECG) analysis are RED and GREEN.

# 29

# **Importing Lens and Coating Data**

The following section describes how lens data from other design packages or from lens catalogues can be imported. Currently supported are optical design packages from CODE-V, ZEMAX, OSLO, MODAS, ATMOS, WinLens, as well as designs from standard catalogue lenses. It is, however, important to note that due to constant improvements in software development, only a subset of the individual design packages will be successfully translated. OpTaliX attempts to recognize a maximum amount of commands and features stored in external lens design files.

Import is accomplished by the generic "IMP" command with optional parameters.

# **29.1** Import of CODE-V Sequential Files

The import of CODE-V sequential files is accomplished by:

imp. co.cl.co.dou	Import CODE-V sequential file from file_spec. Example:
Tub sedicoder	imp seg c·/codev/dblgauss seg
file_spec	imp beg e./eodev/abigaabb.beg

# 29.2 Import of ZEMAX Files

From the command line:

	Import ZEMAX file from file_spec. The correct file
	extension . ZMX must be added
imp zmx zemax file	Example:
file_spec	<pre>imp zmx file c:/zmx_examples/dblgauss.zmx</pre>

From the menu, select

FILE / IMPORT / ZEMAX which opens a file selection box.

# 29.3 Import of OSLO Files

From the command line :

<pre>imp osl[o] file file_spec</pre>	Import Oslo file from file_spec. The correct file extension .LEN must be added
	Example:
	imp oslo file c:/oslo_examples/dbigauss.len

from the menu, select:

FILE / IMPORT / OSLO which opens a file selection box.

# 29.4 Import of MODAS Files

MODAS (Modern Optical Design and Analysis Software) is an amateur program, written by Ivan Krastev.

	Import Modas file from file_spec. The correct file extension
imp mod[as]as	.dsg must be added. Example:
file file_spec	<pre>imp modas file c:/modas_examples/cassegr.dsg</pre>

from the menu, select:

FILE / IMPORT / MODAS which opens a file selection box.

Note on aspheric surfaces: MODAS uses an additional quadratic term  $A_2h^2$  to the aspheric definition in Eq. 8.1 (page 71). This term describes a parabola, which is equivalently modeled by the conic constant K = -1. Since MODAS only allows either a pure conic surface or a higher-order asphere, but not both simultaneously, a simple relation for converting coefficients can be established:

$$c = 2 \cdot A_2 \tag{29.1}$$

Thus, on import MODAS aspheres, the conic constant K will be set to -1 (parabola) and the curvature is set to c. The inverse procedure is applied on export to MODAS.

# 29.5 Import of ATMOS Files

ATMOS is an amateur program, written by Massimo Riccardi, Italy.

	Import Atmos file from file_spec. The correct file extension .atm
<pre>imp atm[os] file file_spec</pre>	must be added
	Example:
	<pre>imp atmos file c:/modas_examples/cassegr.atm</pre>

from the menu, select:

FILE / IMPORT / ATMOS which opens a file selection box.

# **29.6** Import of WinLens Files

From the command line:

	Import WinLens file from file_spec. The correct file exten-
<pre>imp winl[ens] file file_spec</pre>	sion .spd must be added Example:
	<pre>imp winl file c:/examples/dblgauss.spd</pre>

From the menu, select

FILE / IMPORT / WinLens which opens a file selection box.

# 29.7 Import of Accos Files

From the command line:

imp acc[os]	Import lens system in Accos format. This command opens a di-
	alog box for selecting optical designs from library files. Accos
	stores lenses in lens libraries of roughly 2 Mbyte each. Each
	library may contain 98 lenses, called lens library blocks, plus a
	lens in working storage. Lenses have limits imposed in terms
	of number of surfaces, clear apertures etc.

From the menu, select

FILE / IMPORT / Accos which opens a file selection box.

# 29.8 Import of Sigma Files from Kidger-Optics

From the command line:

	Import Kidger-Optics Sigma file from file_spec. The fol-
	lowing formats are supported
	Sigma-PC, which is identified by the file extension . DAT
imp sigma sigmapc	Sigma 2000, which is identified by file extension . LEN
file file_spec	Examples:
	<pre>imp sigma file c:/examples/dblgauss.len</pre>
	<pre>imp sigmapc file c:/examples/dblgauss.dat</pre>

From the menu, select

FILE / IMPORT / Kidger Optics / Sigma which opens a file selection box.

# 29.9 Import Coatings from "The Essential MacLeod" Thin-Film Package

From the command line:

	Import coating design file in the "Essential MacLeod" format
imp macl filo	from file_spec.
file spec	Example:
	<pre>imp macl file c:/ar_coat.dds</pre>

From the menu, select

COATINGS / IMPORT / MacLeod which opens a file selection box.

# **29.10** Import Coatings from the "TFCalc" Thin-Film Package

From the command line:

	Import coating design file in the "TFCalc" format from
<pre>imp tfc file file_spec</pre>	file_spec. Example:
	<pre>imp tfc file c:/ar_coat.dds</pre>

From the menu, select

COATINGS / IMPORT / TFCalc which opens a file selection box.

# 29.11 Import Coatings from the "Optilayer" Thin-Film Package

From the command line:

	Import coating design file in the "Optilayer" format from
imp opti file	file_spec.
	Example:
1116-5666	<pre>imp opti file c:/ar_coat.ods</pre>

From the menu, select

COATINGS / IMPORT / Optilayer which opens a file selection box.

# 29.12 Import from Lens Catalogs

OpTaliX has the capability to read and extract lens systems from lens catalogues of various manufacturers and distributers (e.g. Melles Griot, Newport, Linos, etc).

From the main menu, extract a particular lens from a catalogue by

*FILE / IMPORT / Catalogues*, or *FILE / Catalog Lenses* 

📢 Import Lens from Catalogue	2	
Select Catalogue	Select Item	
Corning CVI-Laser Ealing Edmund Optics ESCO Geltech ISP Optics JML LightPath Linos Photonics Melles Griot Newport Corp. NSG Optics for Research	01LAL007       Laser-Grade Achromat - Standard       F=25,0000         01LAL009       Laser-Grade Achromat - Standard       F=30,0000         01LAL011       Laser-Grade Achromat - Standard       F=40,0000         01LAL013       Laser-Grade Achromat - Standard       F=50,0000         01LAL015       Laser-Grade Achromat - Standard       F=50,0000         01LAL015       Laser-Grade Achromat - Standard       F=75,0000         01LAL017       Laser-Grade Achromat - Standard       F=100,0000         01LAL401       Laser-Grade Achromat - Lead-free       F=10,0000         01LAL403       Laser-Grade Achromat - Lead-free       F=20,0000         01LAL403       Laser-Grade Achromat - Lead-free       F=25,0000         01LAL403       Laser-Grade Achromat - Lead-free       F=20,0000         01LAL404       Laser-Grade Achromat - Lead-free       F=20,0000         01LAL407       Laser-Grade Achromat - Lead-free       F=20,0000         01LAL401       Laser-Grade Achromat - Lead-free       F=30,0000         01LAL411       Laser-Grade Achromat - Lead-free       F=40,0000         01LAL411       Laser-Grade Achromat - Lead-free       F=50,0000         01LAL413       Laser-Grade Achromat - Lead-free       F=50,0000         01LAL415       Laser-Grade Achromat - Le	D=12.0( D=12.0( D=15.0( D=25.0( D=25.0( D=40.( D=40.( D=12.0 D=12.0 D=12.0 D=12.0 D=15.0 D=20.0
Loading Method Make a new system Insert BEFORE surface Filter EFL Diam 0.00 -		$\geq$
	Cancel DK	

Figure 29.1: Dialog for selecting and importing lenses from vendor catalogs.

From the command line, extract a file from a catalogue by the command: imp cat [cat\_ident code\_string] [sk] The lens is identified by code\_string in the catalogue described by cat\_ident. If neither cat\_ident nor code\_no is specified at the command line, a dialog box is opened to select vendor and code number. If surface sk is provided, the system is inserted to the existing system **before** surface sk, otherwise a new system is built.

cat\_ident is a short form of the vendor name, specify one of (only the first three respectively four characters are significant):

- ARCH Archer OpTx COHE Coherent Scientific CORN Corning
- CVI CVI-Laser
- EAL Ealing
- EDMU Edmund Optics
- ESCO Esco
- ${\tt GELT} \quad Geltech$
- ISP ISP-Optics
- JML JML
- LPT LightPath Inc.
- LINO Linos Photonics
- MELL Melles Griot
- NEWP Newport Corporation
- NSG Nippon Sheet Company
- OFR Optics for Research
- OPTO OptoSigma
- PHIL Philips
- QUAN Quantum
- ROLY Rolyn Optics
- ROSS Ross Optical
- SIGM Sigma-Koki, Japan
- SPEC Special Optics
- THOR ThorLabs
- 3M 3M Precision Optics

### Examples:

imp cat melles lpx027
imp cat mell lpx027
imp cat ! invokes a dialog box
imp cat linos 322286 s4 ! inserts Linos achromat before surface 4.

# 30

# **Exporting Lens Data**

The following section describes how OpTaliX lens data can be exported to other optical design packages. It is important to note that due to constant improvements in software development, only a subset of the options respectively commands provided by the individual design packages can be successfully translated. However, OpTaliX attempts to recognize a maximum amount of commands and features provided by other packages. The capabilities of OpTaliX for converting features are constantly improved.

Export is accomplished by the generic "EXP" command with additional parameters.

## **30.1 Export to Code V**

From the command line :

exp seq file file_spec	Export to CODE-V sequential file. Example: exp seq
	c:/temp/dblgauss.seq
wrl file_spec	Writes lens data to Code V sequential (.seq) file.

From the menu, select : FILE / EXPORT / CODE-V which opens a file selection box.

# **30.2 Export to ZEMAX**

From the command line:

exp zmx file file_spec	Export to Zemax file . The correct file extension . ZMX must be added
	exp zmx file c:/temp/dblgauss.zmx

From the menu, select FILE / EXPORT / ZEMAX which opens a file selection box.

# **30.3 Export to OSLO**

From the command line :

	Export to Oslo file. The correct file extension .LEN
	must be added
exp osijosio ille	Example:
IIIe_spec	exp oslo file c:/temp/dblgauss.len

All glasses used in the system are written to a private glass catalogue file in a format expected by OSLO. If required, the glasses contained in the file <code>\optalix\temp\oslo\_private.glc</code> can be merged with the OSLO private catalogue using an ASCII text editor.

From the menu, select:

FILE / EXPORT / OSLO which opens a file selection box.

By default, OpTaliX also exports glass data to a separate file being compatible with the OSLO private glass catalog. This file is found at  $i\temp\oslo_private.glc$ . This feature is particularly useful for glasses not found in OSLO, for glasses with n,  $\nu$  offsets and for exact transfer of fictitious glasses. These glasses may then copied/added to your OSLO private glass catalogue.

# **30.4 Export to ASAP**

ASAP, optical modelling software, is a software package distributed by Breault Research Organization [5].

	Export to ASAP. The correct file extension . INR must be added. The file specification (path + file name) must be enclosed in quotes if file_spec contains blank characters or other special characters (-, &). The optional parameter RAY exports ray sets corresponding to the field points defined in the system.
exp asap file file_spec [RAY]	Examples: exp asap fil c:/temp/dblgauss.inr exp asap file c:/temp/dblgauss.inr RAY ! ex- ports rays as well
	contains special characters

## **30.4.1** Exporting Special Surfaces to ASAP

Special surfaces which do not have an equivalent representation in ASAP must be modelled using the USERFUNC option. This requires definition of a user-function in the ASAP script.

If special surfaces exist in an optical system OpTaliX adds appropriate commands to the exported ASAP script (\* . INR). For example, an anamorphic surface (AAS) would be exported as

where the corresponding function definition is provided with OpTaliX and is found in the directory  $illowide transformation for the maximum of the the example given above you may wish to copy the "BICONIC_FUNC.INR" file to your ASAP working directory.$ 

# **30.5 Export to MODAS**

MODAS (Modern Optical Design and Analysis Software) is an amateur program, written by Ivan Krastev. From the command line :

	Export to Modas file format. The correct file extension				
exp mod modas file	.dsg must be added				
	Example:				
TITE-Spec	<pre>exp modas file c:/temp/cassegr.dsg</pre>				

from the menu, select:

*FILE / EXPORT / MODAS* which opens a file selection box. See also the notes in section 29.4 on exporting aspheres.

# **30.6 Export to ATMOS**

ATMOS is an amateur program, written by Massimo Riccardi. From the command line :

	Export to Atmos file format. The correct file extension
exp atm atmos file	.atm must be added
	Example:
lile_spec	exp atmos file c:/temp/cassegr.atm

from the menu, select:

FILE / EXPORT / ATMOS which opens a file selection box.

# **30.7** Export of Wavefront to ABERRATOR

"Aberrator"[1] is a freeware program written by Cor Berrevoets, Netherlands, that generates startesting images in order to show the effects of aberrations. It computes the diffraction PSF from the exported wavefront and displays it as a gray-coded bitmap, in a similar way as obtained in OpTaliX via the PSF DF or PSF FF commands. At the command line enter :

exp wav [fi wi] file file_spec	Export wavefront to "Aberrator" file format. The correct				
	file extension . opd must be added				
	Example:				
	exp wav file c:/temp/wavefront.opd				

from the menu, select:

FILE / EXPORT / Wavefront to Aberrator which opens a file selection box.

# **30.8** Export to Persistence of Vision (POV)

"Persistence of Vision" (POV) is a freeware general rendering and animation software which may be used to create almost photo-realistic images of the optical design.

From the command line:

	Export to Persistence of Vision (POV) file . The correct file			
	extension ". POV" must be added. In absence of path infor-			
	mation, the file will be stored in the current working directory.			
exp pov file file_spec	The optional parameter ray exports the user defined rays as			
[ray]	defined by the SET FAN command.			
	Example:			
	exp pov file c:/pov_examples/dblgauss.pov			

From the menu, select: *FILE / EXPORT /POV* which opens a file dialog box.

In order to write files in the POV-format, it is not required to have POV installed on the same machine. However, for testing purposes and to check whether the optical system has been successfully transferred, a working installation of POV is recommended. See also section 10.1, page 189 on how to interface OpTaliX with POV.

Note: A similar mechanism is used in the rendering option of the lens draw section (see REN command). The major difference is that the renderer (POV) is directly called.

# **30.9 Export to IGES**

Exchanges optical surface models as 3D geometry to other computer-aided design (CAD) programs in the IGES 5.3 (Initial Graphics Exchange Specification) format. Exported models may include trimmed surfaces, rays, apertures and lens edges. A pure wire-frame option is also available.

	Export optical system to IGES. The correct file extension				
	.igs must be added. IGES output is controlled by the op-				
	tional parameters:				
	sur export surfaces (=default)				
	ray export rays as defined in the VIE				
	option				
own igg four row wir one	wir export a wire-frame model (sim-				
<pre>edg all] [sij sk] [zk] [?] file file_spec</pre>	ilar to 3D lens view)				
	ape export aperture bounds				
	edg export lens edges				
	all export all (surfaces + rays +				
	edges + wire-frame)				
	Absence of any option defaults to SUR, for all surfaces, at				
	zoom position 1. Examples:				
	exp igs sur ray file c:/temp/test.igs				
	exp igs ape ?				

## **30.9.1** Illustration of IGES Export Options

This section illustrates the export options SUR, RAY and WIR. Note that the colour rendering may vary, depending on your preferred CAD system.

Figure 30.1: IGES export with wire frame only option (Command: 'exp igs wir')

Figure 30.2: IGES export with surface only option (Command: 'exp igs sur')

Figure 30.3: IGES export with surface and ray only options (Command: 'exp igs sur ray', alternatively use exp igs all)

## **30.9.2** Supported IGES Entities

Entity Type Number	Description	Comment
102	Composite curve	
106	Copious data	Form number 12
108	Plane	
110	Line	
112	Parametric spline curve	
114	Parametric spline surface	
120	Surface of revolution	
124	Transformation Matrix	
128	Parametric B-Spline surface	In preparation
142	Curve on parametric surface	
144	Trimmed parametric surface	

## **30.9.3 IGES Export Limitations**

OpTaliX tries to export as many construction features as possible. However, not all properties could be supported in the current version.

• Non-rotationally symmetric surfaces (such as cylinders, toroids or free-form surfaces) are represented by a grid of curves, instead of a continuous parametric surface representation as in rotationally symmetric surfaces.

- Only circular and rectangular surface apertures are supported. Elliptical and polygon apertures will be added in future releases.
- Export of edges is not supported for elliptical or polygon apertures, and for decentered circular apertures.

## 30.9.4 IGES Trouble Shooting

Converting CAD data is a complex process. The quality of the translation depends on the diligence and understanding of the people involved, on both sides of the exchange.

IGES is a standard almost 20 years old, now in its sixth revision. Its successor is known as STEP (Standard for Exchange of Product information). After release 5.1, IGES was supposed to metamorphose gracefully into STEP 1.0. But it hasn't worked out that way. There are simply too many active IGES users and too few STEP users to shut IGES down completely. This is also the reason why OpTaliX offers an IGES interface.

The major problem with IGES is that it mostly creates problems! At least it does not work perfectly, not for all people, and not all the time. A complete list of problems people encounter with 3D IGES files would fill a book, so let us identify the general categories of problems.

- The 'law' written into the IGES specification is subject to interpretation and it contains loopholes. Over the years, different brands of CAD companies have interpreted different parts of IGES in uniquely different ways, creating incompatibilities and "flavours".
- There is a large number of ways IGES data can be written. For example, users can export analytic surfaces such as cones and planes as spline surfaces before exporting. Some CAD systems would prefer the the analytic version, others the Spline representation. Also, a cubic spline may be presented as IGES entity 112 or 126 or even as a polyline of points (entity 106).
- Tolerances, accuracy, and resolution: The IGES problem this creates is when IGES files are moved between two CAD/CAM products using different accuracies. Moving a coarse toleranced IGES file to a fine toleranced system produces curves that don't close and surfaces that have gaps and overlaps. Moving a fine toleranced IGES to a coarse toleranced system loses detail for the opposite reason.
- Entity 108 (cubic spline) may not be supported by your preferred CAD system. This entity is often used (also by OpTaliX) for general (2D or non-rotationally symmetric) surfaces.
- Much trouble is caused with raw spline curve and surface geometry (entities 126 and 128).
- Pay special attention to trimmed surfaces (IGES entity 144). The trimming curves can be misplaced or are self intersecting.
- Be sure to look for curves or lines that extend beyond their required limits.
- In general, check if the entities written by OpTaliX (see section 30.9.2, page 501) are suported (recognized) by your CAD system.

# **30.10** Export to Microsoft<sup>TM</sup> Excel File

Certain output data can be exported to a format compatible with Microsoft  $Excel^{TM}$ . This is not a general output switch (such that it would be available on *any* text output) because it is only available for a particular set of data which can be provided as gridded (or tabulated) data.

The ability to provide calculation data in Excel format is based on the installation of Microsoft's ODBC drivers. This requirement is fulfilled if Excel is installed on the target system. Alternatively, it is sufficient to install the "Microsoft Access Database Engine 2010 Redistributable" which may be downloaded from the Microsoft website free of charge, for example

http://www.microsoft.com/en-us/download/details.aspx?displaylang=en&id=13255.

Since export to Excel is based on the ODBC drivers, the export is also bound by the limitations inherent to the ODBC interface. These are namely,

- New data can only be added. It is not possible to address specific cells.
- Only data types NUMBER, DATETIME, TEXT, CURRENCY and LOGICAL are supported. It is not possible to transfer arithmetic equations or other formats.
- Text formatting (colour, font, etc.) is not possible.
- The maximum length of column names is limited to 63 characters.

Exported data from OpTaliX is found in a sheet labelled "Data" as shown in the figure below (Fig. 30.4):

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	A1	+0	<i>fx</i> "T	HI_S5_'						Y
	A	В	С	D	1	E	1	F	G	T_
1	THI_S5_' ]"	THI_S10'	'THI_S15'	'EFL'		'OAL'	'SPD_	F1'		
2	1	56.472014	1.1249861	5.903	314	121.5	0.00	375945		
3	3	54.371534	1.2254662	6.2521	439	121.5	0.003	625637		
4	5	52.265173	1.3318265	6.6326	683	121.5	0.003	500935		
5	7	50.151508	1.4454916	7.049	124	121.5	0.003	402812		-
6	9	48.031848	1.5651525	7.5054	566	121.5	0.00	332214		
7	11	45.905089	1.6919111	8.0070	724	121.5	0.003	270615		
8	13	43.769381	1.8276193	8.5605	901	121.5	0.003	274781		
9	15	41.624453	1.9725468	9.173	095	121.5	0.003	344609		
10	17	39.469358	2.1276419	9.8531	928	121.5	0.003	494507		
11	19	37.303017	2.2939834	10.611	098	121.5	0.003	742044		
14 4 1	N Data	2 Como	~ /70000 /		1	4		******	+	D
Bereit	t				Um	回四 10	0%		0 4	2

Figure 30.4: Example export to  $Excel^{TM}$  from a zoom CAM calculation.
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## **Examples Library**

OpTaliX provides an extensive library of starting designs, comprising more than 500 designs from publications and patent literature. This also includes the complete libraries from Arthur Cox, Warren Smith, and from the Wiley "Handbook of Optical Design, Vol 4".

The example designs are stored during installation of OpTaliX in the folder

\$i\examples

In the program, the example files can be browsed from the command line

 EXAMP
 Invokes a dialog box for selecting various example designs.

or from the main menu

(( <b>%</b> O	pTali	X-Pro	6.98	D:\optalix\exa	mples\Misc
File	List	Edit	Display	Geom.Analysis	Diffr.Analys
N	ew				Ctrl+N
0	pen				Ctrl+O
S	ave				Ctrl+S
S	Save As				
Print					
Examples Library					
Export •					
In	nport				•
Pi	refere	nces .			Ctrl+P

Figure 31.1: Menu entry for selecting the Examples Library

A typical dialog box is shown in Fig. 31. Select the design category and the design file in the tree-view to the left. Pressing OK loads the selected design. CANCEL resumes to the previously loaded design.



Figure 31.2: Selecting an example design from the library

## **File Formats**

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All files used or created by OpTaliX are plain ASCII files which may be edited by any text editor.

## **32.1** *OpTaliX* **Configuration File "optix.cfg"**

The OpTaliX configuration file "optix.cfg" stores a number of settings (mainly path information) which are used during each session. The file must reside in the OpTaliX installation (home) directory. The information is stored in free-form ASCII format and thus, may be read and edited by any text editor.

All entries are separated by at least one blank, multiple blanks as separator are permitted. The exclamation character "!" is identified as comment.

Qualifiers and parameters are separated by the equal " = " character. The qualifiers and its corresponding parameters are:

RENDER = path_string	Path to an external rendering program for generation of shaded
	perspective 3-dimensional views of the lens layout. To use
	this feature, the official version of the "Persistance of Vision"
	(POV) raytracer must be installed separately.
HTML = path+exe_string	Path to an external HTML browser. This path is mandatory
	to have access to the online help manual. This entry will be
	created during installation. Modify it if a different browser
	shall be used.
GLASSES = path_string	Path to glass catalogues. This entry is commented by default
	and should not be modified (except if you exactly know what
	you are doing).
COATINGS = path_string	Path to coatings files.
TEMP = path_string	Path to temporary working directory
MACRO = path_string	Path to macro files and user defined graphics definitions.
SAVDEFAULTONEXIT = int	Save the current system on program exit. int is an integer
	number. $0 = don't$ save, $1 = save$ .
SAVWINONEXIT = int	Save window settings (position, size) on program exit, 0=no,
	1=yes
TEXTFOREGR = int	Put text output window to foreground each time new output is
	generated, 0=no, 1=yes

#### An example of an OpTaliX configuration file is:

```
! Optix configuration file
```

```
! Entries must be separated at least by one blank character
```

```
! Characters are case insensitive
```

```
! Path names containing blanks must be enclosed in quote character (")
!
HTML =
RENDER = "f:\pov31a\bin\pvengine.exe"
!
! Uncomment and edit the following lines only if you wish a
! different search path for glasses, coatings or temp.
!
! GLASSES = "e:\optix\GLASSES\"
! COATINGS = "e:\optix\coatings\"
! TEMP = "e:\optix\temp\"
```

As can be seen from the example above, some qualifiers (GLASSES, COATINGS, ..) are commented. The default paths are used instead (i.e. below the OpTaliX installation directory).

## 32.2 Lens Prescription Format ".otx"

The lens data are stored in standard unformatted ASCII file with the extension ".otx". In each line, the lens prescription parameters are identified by a keyword. All entries are separated at least by one blank, multiple blanks as separator are permitted. The exclamation character "!" is identified as comment.

The keywords and the possible (allowed) parameters are described in alphabetical order in the following table. The type of the variables is indicated by "int" for an integer value, "real\_val" for a real value and "char" for a character string.

	Asymmetric aperture (for lens cross sectional plot only)
	int = 0 : full surface aperture is plotted
AAP INC	int = 1 : only the section used by the light beam is
	plotted
ADE real_val	Surface tilt around X-axis, in degree
AFO int	Afocal switch, int = 1: system is afocal.
	Aperture definition
	int = pupil number (default = 1)
	val1 = semi aperture in X
	val2 = semi aperture in Y
	val3 = X-offset of aperture from surface vertex
	val4 = Y-offset of aperture from surface vertex
APE int vall val2	val5 = rotation angle (in degree)
val3 val4 val5 int2	int2 = pupil type (1=circular, 2=rectangular, 3=elliptical,
int3 int4	4=polygon)
	int3 = logical operator (0=base pupil, 1= logical and, 2=logical
	or)
	int4 = transmission properties (0=inside, 1=obstruct, 2=hole)
	Circular aperture
	int = pupil number (default = 1)
	val1 = semi aperture in Y
APEC int vall int2	int2 = logical operator (0=base pupil, 1= logical and, 2=logical
1nt3	or)
	int3 = transmission properties (0=inside, 1=obstruct, 2=hole)
	continued on next page

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AFR real_val	Autofocus spatial frequency in line pairs. This is the spatial
	frequency, at which the MTF-autofocus is determined.
	Aspheric coefficients,
ASP val1 val2	val1 = conic constant
val7	val2 val7 = polynomial coefficients
ARX real_val	Array X-spacing of channels
ARY real_val	Array Y-spacing of channels
ARXO real_val	Array X-offset
ARYO real_val	Array Y-offset
AXG real_val	Tolerance: axial linear gradient
BDE real_val	Surface tilt around Y-axis, in degree
BIR val1 val11	Refractive index of birefringent material
CDE real_val	Surface tilt around Z-axis, in degree
COA string	File name of coating, attached to current surface
COM string	Comment per surface
CON string	Optimization constraints
CTV icoeff real_val	Coating thickness variation coefficient, icoeff is the coeffi-
	cient number between 1 and 5, real contains the coefficient.
CUX real_val	X-curvature
CUY real_val	Y-curvature
DEF real_val	Defocus of real image plane from paraxial focus
DLA real_val	Tolerance: alpha tilt (about X-axis)
DLB real_val	Tolerance: beta tilt (about Y-axis)
DLG real_val	Tolerance: gamma tilt (about Z-axis)
DLF real_val	Tolerance: Test plate fit in fringes
DLN real_val	Tolerance: index of refraction
DLR real_val	Tolerance: absolute radius in mm
DLT real_val	Tolerance: axial thickness in mm
DLV real_val	Tolerance: dispersion (Abbe number) in %
DLX real_val	Tolerance: X-decenter
DLY real_val	Tolerance: Y-decenter
DLZ real_val	Tolerance: Z-decenter
DTR real_val	Tolerance: reference thickness in mm
DNO real_val	$\Delta n$ - Offset
DVO real_val	$\Delta \nu$ - Offset
EPD real_val	Entrance pupil diameter
EXC real_val	Linear expansion coefficient in $10^{-6}$ units
FACT i_active1	Field activation. A particular field point may be excluded from
i_active2	analysis, i.e. it is not active. i_active is an integer number
	(0 = inactive, 1 = active) and counts from 1 to the maximum
	number of fields (defined by FLDX and FLDY)
	Fixed aperture height,
FH int	int=0 : aperture does not limit/truncate light beam
	int = 1 : aperture defines/truncates light beam
FIBS string	Specify source fiber by product (e.g. by manufacturers type
	number).
	continued on next page

continued from previous page	1		
FIBR string	Specify receiving fiber by product (e.g. by manufacturers type		
	number).		
FILE string	File name (optional)		
FNO real_val	F-Number		
FLDX val1 val11	Field coordinate in X.		
FLDY val1 val11	Field coordinate in Y.		
	Alternative form of specifying field points. Use either		
	FLDX/FLDY or FLD entry.		
	int = field number		
FLD int x_field	x_field = X-field coordinate, meaning depends on FTYP		
y_field weight active	y_field = Y-field coordinate, meaning depends on FTYP		
	weight = field weight		
	active = $0/1$ , defines whether field point is used in analysis.		
	Fresnel narameter		
FRES val1 val2	val1 = X-tilt of fresnel facets		
	val2 = Y-tilt of freshel facets		
FRA alpha tilt	Receiving fiber $\alpha$ -tilt in degree		
FRB beta tilt	Receiving fiber $\beta$ -tilt in degree.		
FRD real val	Ear-field divergence of receiving fiber (in rad)		
FRN1 real val	Receiving fiber index of refraction $n_1$ of core material		
FRN2 real val	Receiving fiber, index of refraction $n_2$ of cladding material		
FRCR real val	Receiving fiber, one radius in mm		
FRR mode radius	Receiving fiber mode-field radius in mm		
FRX x-offset	Receiving fiber, mode note name		
FRY v-offset	Receiving fiber v-offset (in mm)		
FSA alpha tilt	Fiber source $\alpha$ -tilt in degree.		
FSB beta tilt	Fiber source $\beta$ -tilt in degree		
FSD div x div y	Far-field fiber source divergence (in radians) in X- and Y-		
	direction.		
FSN1 real_val	Source fiber, index of refraction $n_1$ of core material		
FSN2 real_val	Source fiber, index of refraction $n_2$ of cladding material		
FSCR real_val	Source fiber, core radius in mm.		
FSR rad_x rad_v	Fiber source radius in X- and Y-direction (in mm).		
FTH f_thick	Fresnel thickness		
	Field type		
	int = 1 : Field coordinates are defined by field angle		
FTYP int	int = $2$ : fields are defined by object coordinates		
	int = 3 : fields are defined by paraxial image coordinates		
	int = 4 : fields are defined by real image coordinates		
FWGT int1 int10	Field weights		
GIC val1 val50	Gradient index coefficients. The number of coefficients is de- fined by NGIC.		
GIS real_val	Gradient index step, the integration distance in gradient index		
	material		
GIT string	Gradient index type (e.g. SEL, AXG, LPT, URN)		
GLA string	Glass name (up to 10 characters)		
	continued on next page		
	continued on none page		

r

continued from previous page			
GL1 string	Glass name, defines material left to surface (only applicable for		
	NSS)		
GL2 string	Glass name, defines material right to surface (only applicable		
	for NSS)		
GRO real_val	Grating order		
GRX real_val	Grating constant in X-direction, applicable only for a straight-		
	line ruled grating		
GRY real_val	Grating constant in Y-direction, applicable only for a straight-		
	line ruled grating		
	Gradient profile tilt/decenter		
	val1 val3 : X,Y and Z decenter of gradient profile		
GIILI VALI VALO	val4 val6 : $\alpha, \beta, \gamma$ - tilts around X-, Y-, and Z-axis respec-		
	tively		
GZO real_val	Gradient Z-Offset of profile definition from surface vertex (ap-		
	plicable only for axial profiles from LightPath).		
HWL real_val	Hologram design wavelength, in microns		
HCO icoeff real_val	Hologram coefficient, icoeff is the coefficient number be-		
	tween 1 and 28.		
HOM real_val	Tolerance: index homogeneity		
HOR order	Hologram diffraction order		
HOT int	Hologram type, int = $0$ for a straight-line ruled grating, $1$ for a		
	symmetrical phase function, 2 for an asymmetrical (2d) phase		
	function		
HX1 obj_source_x	X-coordinate of object point source for holographic surface.		
HY1 obj_source_y	Y-coordinate of object point source for holographic surface.		
HZ1 obj_source_z	Z-coordinate of object point source for holographic surface.		
HX2 ref_source_x	X-coordinate of reference point source for holographic surface.		
HY2 ref_source_y	Y-coordinate of reference point source for holographic surface.		
HZ2 ref_source_y	Z-coordinate of reference point source for holographic surface.		
IRR real_val	Tolerance: irregularity in fringes		
KLDR	For internal use only, not required (controls plot appearance)		
LINK int1 int2 int3	Link(pickup) surface (curvature, thickness,tilt,material)		
int4			
	Lens module (ideal lens)		
LMOD val1 val5	val1 = focal length		
	val2 val5 : not yet defined		
MZ VAL	quanty factor <i>M</i> <sup>-</sup>		
MER real_val	Mada models assume "acting" much any formation		
MPRS string	mode profile. STER for stars index, ETT, for stars in for the STE		
	node prome, STE for step-index, FTL for user defined profile		
MDDD at a '	Ioaded from file.		
MPRK string	vioue profile, receiver. "string" may be any of GAU for Gaus-		
	sian mode profile, STE for step-index, F1L for user defined		
	prome loaded from file.		
MXH int	Maximum hits (of rays at a non-sequential surface).		
NA real_val	Numerical aperture, in image space		
NAO real_val	Numerical aperture, in object space		
	continued on next page		

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NGIC int	Number of GRIN-coefficients
NSS int	Non-sequential surface
	int = 0 : sequential, int = 1 : NSS-surface
NTOF int	Number of tolerance functions.
OSP spectrum_name	Optical spectrum. The spectrum names are defined in the file
	osp.dat
PCO real_val	Partial dispersion P(C,s)-Offset
PGO real_val	Partial dispersion P(g,F)-Offset
PLSC	For internal use only. (Plot scaling)
	Polarization switch
POL int	int = 0: polarization is ignored
	int = 1 : polarization is taken into account.
	Polarization state of input wave I
POL1 val_x val_v	val_x = X-amplitude
valph	$val_y = Y$ -amplitude
	val_ph = Phase
	Polarization state of input wave 2
POL2 val_x val_y	$val_x = x$ -amplitude
val_ph	$val_y = Y$ -amplitude
	val_ph = Phase
PRI VAII VAIII	Private glass. vali vali i are the indices of refraction at the
	wavelengths defined in WL.
PRE real_val	Pressure in mmHg
PUI real_val	Pupil intensity (to be used in combination with PUX, PUY).
PUX real_val	Relative X-coordinate (refered to entrance pupil radius) for PUI
	value
PUY real_val	Relative Y-coordinate (refered to entrance pupil radius) for PUI
	value
RAG real_val	Tolerance: radial quadratic gradient
	User defined ray coordinates at entrance pupil.
	string = ray type
RAY string val1	val1 = X-coordinate of ray
val5	val2 = Y-coordinate
	val3 val5 = X, Y, Z direction cosines
	Kay aiming method
RAIM int	int = 0 : rays are aimed to paraxial entrance pupil (no iteration)
	int = 1: rays are aimed to real stop, iteration is performed.
	int = 2: telecentric ray aiming
RAII real_val	tion to the need store surface.
	non to the real stop surface.
RCX VAL	Radius of curvature of wavefront at object plane in x-direction
RCY VAL	Radius of curvature of wavefront at object plane in y-direction
REF int	Reference wavelength number
REM int string	Remarks, "int" is the surface number, "string" containes the
	remark text (up to 80 characters)
	continued on next page

continued from previous page	
	Surface reference
	iref: reference surface
	val1: reference thickness (THR)
SREF iref vall	val2 val4 : X,Y and Z decenter wrt. reference sur-
val7	face iref
	val5 val7 : $\alpha, \beta, \gamma$ - tilts around X-, Y-, and Z-axis
	respectively
SPLR icoeff rad	Radial spline deformation. icoeff is the running num-
z_deform	ber of the deformation point, rad is the radial component,
	z_deform is the deformation (in mm).
SUR int	Surface identifier. Increments the surface counter.
SUT string	Surface type
STO	Surface is aperture stop
TEM real_val	Temperature in degree Celsius
TGR int	Transformation grid size
THI real_val	Thickness (axial separation) to next surface.
	Surface tilt/decenter
	val1 val3 : X,Y and Z decenter
TILT VALL VAL6	val4 val6 : $\alpha, \beta, \gamma$ - tilts around X-, Y-, and Z-axis respec-
	tively
TLM int	Tilt mode
TOLC fkn_tol string	fkn_tol = limit on tolerance criterium, string = Tolerance
	criterium string
	Tolerance compensation method.
TOCM int	int = 0: no compensator
	int = 1: back focus
	int = 2 : use setting in optimization.
TOPM int	Compute plus/minus tolerance sensitivity $(0 = no, 1 = yes)$ .
	Transmission switch
TRA int	int = 0: transmission is ignored
VEDS roal wal	int = 1 : transmission is taken into account.
	Ontimization variables
	Zoom variables for optimization
WI. val1 val11	Wavelengths in micron
WEX val	Waist radius in X-direction given in mm
WRY val	Waist radius in Y-direction, given in mm
WTW intl intl	Wavelength weight integer numbers between 0 and 100
XDE real val	Surface X-Decenter
VDE real val	Surface X-Decenter
ZDE real val	Surface 7-Decenter
700	Zoom parameter string
ZPOS int	Number of zoom positions
ZRN val1 val40	Zernike coefficients
ZWX val	Location of beam waist relative to object plane in x-direction
ZWX VAL	Location of beam waist relative to object plane in x direction
LWI VAL	Location of beam waist relative to object plane in y-unection

## 32.3 Multilayer File Format ".otc"

Multilayer coatings are typically stored in the directory i/coatings where i is the installation directory (i.e. where the OpTaliX executable resides). It is, however, possible to specify a different coatings directory by modification of the COATING entry in the "optix.cfg" file.

The coating prescription is stored in standard unformatted ASCII file with the extension ".OTC". In each line, the coating parameter is identified by a keyword. The keywords and the allowed parameters are described as follows:

VEDC	Version number of $OnTali X$ which arouted the coating file
	Comment string england in spectrum media
COM string	Comment string, enclosed in quotation marks, e.g. COM
	"AR-Coating for visible". The comment string may be
	up to 256 characters.
NLY real_val	Number of layers (excluding top and bottom medium (typically
	air and substrate)
LAMO real_val	reference wavelength, in microns
LAM1 real_val	minimum wavelength, needed for plotting purposes only
LAM2 real_val	maximum wavelength, needed for plotting purposes only
TSMIN TSMAX	Minimum and maximum of transmission plot range. The param-
	eter is between 0 and 1. Required for plotting purposes only.
RSMIN RSMAX	Minimum and maximum of reflection plot range. The parameter
	is between 0 and 1. Required for plotting purposes only.
ANGLE real_val	Incidence angle (in degree). Required for plotting purposes only.
PLOT_S int_val	Plot the S-component. $0 = no, 1 = yes.$
PLOT_T int_val	Plot the T-component. $0 = no, 1 = yes.$
PLOT_A int_val	Plot the A-component (average). $0 = no, 1 = yes$ .
LOG int_val	Select logarithmic display (0=no, 1=yes). Use in conjunction with
	FLOOR.
FLOOR real_val	Floor for logarithmic display. For example FLOOR -3.0 defines
	0.001 as the lowest value displayed in plots.
SHOWTARG int_val	Show refinement targets in transmission/reflection plots (0=no,
	1=yes).
PLOT_COL coll col2	Defines colours of curves in transmission/reflection plots, for S-
col3	, T- and Average components. The colour numbers are integer
	values and are calculated in a 24-bit RGB colour space as red +
	green*256 + blue*256**2.
LAY	Layer number. Increments the layer. Numbering starts with the
	incident medium (layer 1) and ends with the substrate (NLY $+$ 2).
GLA	The layer "glass" (material name). A character string up to 64
	characters is accepted. Blank characters and control characters
	(carriage return, end-of-file, tab, etc.) are not allowed. The glass
	name may be any of the standard catalogue glasses (e.g. BK7).
	If not specified, i.e. the glass name is empty (blank characters),
	the refractive index as defined in the IND command will be used
	instead. A glass (material) name is mandatory if dispersion shall
	be taken into account.
	continued on next page

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OTH	Optical thickness, in wavelength units defined at the reference
	wavelength LAMO. OTH is interpreted in the normal direction to
	the stratified layer.
PTH	Physical thickness, in mm. This is an optional parameter, as the
	thickness of a layer is primarily defined by the optical thickness.
	Only in case optical thickness (OTH) is not specified in the in-
	put file, optical thickness is calculated from the physical thickness
	(PTH).
IND [layer_num]	Complex refractive index. This index will be used for all wave-
	lengths, that is, material dispersion effects are ignored unless a
	glass is specified for this layer. layer_num is optional, because
	the key word LAY alone will increment numbering of the layers.
	layer_num is only written for better readability of the coating
	prescription file (*.otc).
PICKUP i_mat i_thi	Picks material and/or thickness properties from a previous layer.
	i mat is the layer number for material pickups, i thi is the
	layer number for thickness pickups.
PFAC real_val	Packing factor describing layer density. A value between 0 and 1.
	Currently not used.

Normally, thin-film layer materials are defined in the catalogue files coat.asc (for pre-defined catalogue materials) and coatp.asc (privately defined layer materials). The definition of layer materials may be embedded with the coating (multi-layer) prescription file \*.otc. The syntax for describing layer material properties within the coating file is defined in the following table 32.4:

Table 3	32.4:	Embedding	laver	materials	in	coating	files:
10010 0							

	The environment BEGIN MATERIAL / END MATE-
	RIAL defines material properties as part of the coating
	prescription, i.e. material properties (n,k) are embed-
	ded in the the coating file (*.otc). The material name
BEGIN MATERIAL mat_name	mat_name is a string of max. 64 characters wide. The
DATA lam n k	DATA statement describes the triple (lam, n, k), where
	lam is the wavelength (in $\mu m$ ), and (n, k) is the the
DATA Idii II K	complex index of refraction
•••	
END MATERIAL	

#### **Example Coating File:**

```
VERS = 2.82
COM = "Antireflection coating for visible range"
NLY = 4
LAM0 = .5460000
LAM1 = .4000000
LAM2 = .8000000
TSMAX = .0000000e+00
TSMIN = .0000000e+00
RSMAX = .5000000e-01
```

```
RSMIN = .0000000e+00
ANGLE = .0000000e+00
PLOT_S = 1
PLOT T = 1
PLOT A = 1
LAY = 1
  GLA =
  OTH = 0.0000000e+00
  PTH = 0.0000000e+00
  IND = 1.0000000 0.0000000e+00
LAY =
       2
  GLA = mqf2
  OTH = 0.24819737
  PTH = 0.98300005e-04
  IND = 1.3785938 0.0000000e+00
LAY = 3
  GLA =
  OTH = 0.50558242
  PTH = 0.12960001e-03
  IND = 2.1300000 0.0000000e+00
LAY = 4
  GLA =
  OTH = 0.20545055
  PTH = 0.68400003e-04
  IND = 1.6400000 0.0000000e+00
!
BEGIN MATERIAL NewMat
  DATA 0.45 1.50 0.0001
  DATA 0.55 1.48 0.0002
  DATA 0.65 1.46 0.0003
END MATERIAL
```

#### Note:

Keywords and parameters may be separated by an equal sign "=". The separator for multiple parameters in a single line can be a comma "," or at least one blank character. OpTaliX correctly interprets formats like:

IND 1.521 0.0d0 IND = 1.521 0.0d0 IND = 1.521,0.0d0

## 32.4 Zernike Deformation File Format ".zrn"

Reading Zernike coefficients from a file is rather straightforward. The coefficients are stored in a free formatted ASCII file where each line contains the number of the coefficient and the coefficient itself:

```
coeff_no coefficient
```

The entries are separated by at least one blank, multiple blanks as separator are permitted. The exclamation character "!" is identified as comment. An example of a valid Zernike coefficient file is

```
! Zernike coefficients at surface 1
        ! here follows more descriptive text
1       0.0003
```

```
3 1.743E-5

14 0.1 ! this is coefficient no. 14

16 -2.345d-12

! end of Zernickes
```

Coefficients for different surfaces must be stored in different files. The standard file naming convention is the 8.3 DOS standard. Longer file names must be enclosed in parenthesis, e.g.

"this is my file.txt"

### 32.5 Radial Spline Deformation File Format

Reading radial Spline deformation coefficients from a file is rather straightforward. The coefficients are stored in a free formatted ASCII file where each line contains two real numbers:

```
radial_distance deformation
```

where :

radial\_distance is the distance in radial direction of the sample point,

deformation is the deformation at the sample point with respect to the base surface.

The entries are all separated by at least one blank, multiple blanks as separator are permitted. The exclamation character "!" is identified as comment. As an example, a valid Spline deformation file is

```
! Spline deformation at surface 1
        ! here follows more descriptive text
1.234   0.0003
3.5 1.743E-5
4.56      0.1     ! deformation is +0.1mm at 4.56mm radial height
        5.9 -2.345d-12
! end of deformations
```

Coefficients for different surfaces must be stored in different files. The standard file naming convention is the 8.3 DOS standard. Longer file names must be enclosed in parenthesis, e.g.

"this is my file.txt"

## **32.6** Test Plate File Format ".tpl"

Test plate lists (TPL) are stored in unformatted ASCII files. Each test plate radius is stored in a single line which contains four entries:

plate\_ID RADIUS MAX\_DIAM CVCX

where:

PLATE_ID	A unique identification string	
RADIUS	Radius of curvature (in mm)	
MAX_DIAM	Maximum test plate diameter	
	·	continued on next page

continued from previous page	
	Availability of test plate:
CNOV	-1 = only concave radius available
	0 = convex and concave radius available
	1 = only convex radius available

All entries are separated by at least one blank character. Comment lines in a TPL file begin with an "!" (exclamation mark). Each entry is separated by at least one blank character. Tabs are allowed and are interpreted as a single blank character. There is no limit on the number of comment lines.

The first lines of a valid test plate file are:

```
! My Company Inc.
!
10000-1 1.00000 1.96 0
14330-1 1.43220 2.81 0
15679-1 1.56800 3.07 0
20833-1 2.08320 4.08 0
21288-1 2.12880 4.17 0
```

### 32.7 Glass Catalogue File Format ".csv"

Optical glasses from vendor catalogues are stored in standard ASCII files which can be read and modified by any text editor that handles ASCII files properly, such as NOTEPAD. We explicitly discourage use of Windows-Word or any similar word processor for editing glass catalogues.

Data for each glass type are stored in a single line where the parameters are separated by commas ",". Note that this file format is compatible with Microsoft Excel CSV files. Glass catalogue data can easily be imported into Excel, manipulated, and subsequently written to a file with extension ".csv".

The first line is obligatory and must contain the string "!GLASSV3" as the first characters. The rest of the line is not significant.

The second line is obligatory and may contain any arbitrary text. Note that the first and second line are not used in reading glass data.

The third line and all subsequent line lines contain glass parameters, one line for each glass type.

The glass catalogue file is ended by an empty line followed by a carriage return (CR) and line feed (LF) character.

#### **Example file:**

!GLASSV3							
!Manufact	.,Name	,EqName	, (	Code , I	B1 ,	В2	
SCHOTT	,N-BAF3	,S-BAM3	,	583466,	1.34859634E+00,	1.07644240E-01,	
SCHOTT	,N-BAF4	,S-BAM4	,	606437,	1.42056328E+00,	1.02721269E-01,	
SCHOTT	,N-BAF10	,S-BAH10	,	670471 <b>,</b>	1.5851495E+00,	1.4355939E-01,	
SCHOTT	,N-BAF51	,N-BAF51	,	652450 <b>,</b>	1.51503623E+00,	1.53621958E-01,	
SCHOTT	,N-BAF52	,N-BAF52	,	609466,	1.43903433E+00,	9.67046052E-02,	
SCHOTT	,N-BAK1	,S-BAL11	,	573576 <b>,</b>	1.1236566E+00,	3.0927685E-01,	
SCHOTT	,N-BAK2	,S-BAL12	,	540597,	1.0166215E+00,	3.1990305E-01,	

```
SCHOTT ,N-BAK4 ,S-BAL14 , 569560, 1.28834642E+00, 1.32817724E-01, ....
SCHOTT ,N-BALF4 ,H-E-BALF4 , 580539, 1.31004128E+00, 1.42038259E-01, ....
SCHOTT ,N-BALF5 , ,547536, 1.28385965E+00, 7.19300942E-02, ....
....
```

The sequence of glass parameters in each line is as follows:

Data type	Description
Manufacturer	Manufacturer's name. The first three characters are significant.
Glass Name	Glass type name as defined by manufacturer. Limited to 64 characters.
Equivalent name	Name of equivalent glass from alternative manufacturer. Limited to
	64 characters.
Code	MIL code as described in sect A six-digit number.
C1	First dispersion coefficient. The meaning of the coefficient is given by
	the dispersion formula, as shown in sect. $13.1$ and the equation type
	shown below .
C2	Second Dispersion coefficient
C3	Third Dispersion coefficient
C4	4 <sup>th</sup> Dispersion coefficient
C5	5 <sup>th</sup> First Dispersion coefficient
C6	6 <sup>th</sup> First Dispersion coefficient
C7	7 <sup>th</sup> First Dispersion coefficient
C8	8 <sup>th</sup> First Dispersion coefficient
C9	9 <sup>th</sup> First Dispersion coefficient
C10	$10^{th}$ First Dispersion coefficient
	Integer number, describing type of dispersion equation.
	0 = old Schott equation (eq. 13.1),
	1 = Sellmeier equation (eq. 13.2)
	2 = Herzberger equation (eq. 13.8)
	3 = Nikon equation (simple)
	4 = Hartmann equation (eq. 13.9)
	5 = Air (eq. 13.18 - 13.8)
	6 = Sweatt diffractive high index model
	7 = not used
	8 = not used
Equation type	9 = Nikon equation (Extended 3), eq. 13.7
	10 = Extended Sellmeier (Sellmeier 3) eq. 13.3
	11 = Nitrogen
	12 = Cauchy (eq. 13.10)
	13 = Vitron infrared eq.
	14 = Conrady equation (eq. 13.11)
	15 = Handbook of Optics 1 (eq. 13.12)
	16 = Handbook of Optics 2 (eq. 13.13)
	17 = Sellmeier $2$
	18 = Reduced Sellmeier (Sellmeier 4) eq. 13.6
	19 = Sellmeier 5 (eq. 13.4)
Lambda_min	minimum wavelength supported by the dispersion equation.
	continued on next page

continued from previous page	
Lambda_max	maximum wavelength supported by the dispersion equation.
Availability (Lv)	Glass availability. $1 =$ highest melt frequency, $6 =$ lowest melt fre-
	quency, $0 = unknown$ .
D0	dn/dT coefficient 1
D1	dn/dT coefficient 2
D2	dn/dT coefficient 3
EO	dn/dT coefficient 4
E1	dn/dT coefficient 5
LTK	dn/dT coefficient 6, $(\lambda_{TK})$
DRT	thickness for internal transmission ("Reintransmission") data, (mm)
$ au_{2500}$	internal transmission at 2500nm, at DRT
	internal transmission at 2325nm, at DRT
$\tau_{1970}$	internal transmission at 1970nm, at DRT
T1520	internal transmission at 1530nm, at DRT
T1060	internal transmission at 1060nm, at DRT
71060	internal transmission at 700nm at DRT
7700	internal transmission at 660nm at DRT
7660	internal transmission at 620nm at DRT
7620	internal transmission at 520nm, at DPT
7580	internal transmission at 546nm at DRT
7546	internal transmission at 540mm, at DRT
$ au_{500}$	internal transmission at 500nm, at DRT
$ au_{460}$	internal transmission at 460nm, at DRT
$ au_{436}$	internal transmission at 436nm, at DRT
$ au_{420}$	internal transmission at 420nm, at DRT
$ au_{404}$	internal transmission at 404nm, at DRT
$ au_{400}$	internal transmission at 400nm, at DRT
$ au_{390}$	internal transmission at 390nm, at DRT
$ au_{380}$	internal transmission at 380nm, at DRT
$ au_{370}$	internal transmission at 370nm, at DRT
$ au_{365}$	internal transmission at 365nm, at DRT
$ au_{350}$	internal transmission at 350nm, at DRT
$ au_{334}$	internal transmission at 334nm, at DRT
$ au_{320}$	internal transmission at 320nm, at DRT
$ au_{310}$	internal transmission at 310nm, at DRT
$\tau_{300}$	internal transmission at 300nm, at DRT
$ au_{290}$	internal transmission at 290nm, at DRT
$ au_{280}$	internal transmission at 280nm, at DRT
$ au_{270}$	internal transmission at 270nm, at DRT
$ au_{260}$	internal transmission at 260nm, at DRT
$ au_{250}$	internal transmission at 250nm, at DRT
no data	intentionally left blank
no data	intentionally left blank
Chemical constants (CC)	
$\alpha_1$	Linear constant of thermal expansion (CTE), $-30^{\circ}$ C to $+70^{\circ}$ C
$\alpha_2$	Linear constant of thermal expansion (CTE), $+20^{\circ}$ C to $+300^{\circ}$ C
0	Specific density (g/cm <sup>3</sup> )
RelPrice	Relative price ( $BK7 - 1.0$ )
	Kenative price (DK7 – 1.0).

### 32.8 Melt Glass File Format ".ind"

Pairs of wavelength and measured refractive index are stored in a standard ASCII-file with extension ".ind" (required). Each pair is stored in a separate line. Wavelengths must be given in  $\mu m$ . All entries are separated by at least one blank, multiple blanks as separator are permitted. The exclamation character "!" is identified as comment. A typical example of a melt data file is

```
! wavel. index
0.435800 1.825150
0.480000 1.816510
0.486100 1.815500
0.546100 1.807510
0.587600 1.803390
0.643800 1.799020
0.656300 1.786080
!
! Data for Schott Lasfn30, batch no. 123456-1
```

## 32.9 GRIN Dispersion Coefficients File Format

Dispersion data for gradient index (GRIN) materials are stored in the file grindisp.asc in the GLASSES directory. Dispersion coefficients are assigned a name, which can be used by the GDISP command to associate that dispersion characteristics to a surface.

The grindisp.asc file contains blocks of 10 lines each. The file format has the following structure:

```
Dispersion name

min_wavelength max_wavelength

ref_wavelength

K_max L_max

K11 K12 K13 K1K_max

K21 K22 K23 K2K_max

K31 K32 K33 K3K_max

L11 L12 L13 L1L_max

L21 L22 L23 L2L_max

L31 L32 L33 L3L_max
```

Multiple materials may be defined by adding blocks of 10 lines one after the other. Blank lines between the blocks are not permitted.

Note that dispersion coefficients defined by a dispersion name require the glass name GRIN on a surface. Predefined gradient index materials will ignore user defined dispersion coefficients. Currently only profiles from LightPath (LPT) and the general URN (University of Rochester) profile accept these coefficients.

Sample grindisp.asc file containing two dispersion profiles "GLAK" and "GSF":

```
GLAK

0.365 0.725

0.58756

4 1

0.00522664 0.0206983 -0.00450304 0.006873

0.0472841 0.0429402 -0.00724884 -0.0445419

0.988601 0.057962 0.0941671 0.152672

0.0421634
```

```
0.0368588

110

GSF

0.38 2.2

0.58756

6 3

-0.0683636 -0.0323639 -0.0286748 -0.0169163 0.00256909 0.0174719

-0.00109783 0.0334663 0.0388098 0.0370413 0.017429 -0.0405421

0.931075 -0.0306245 -0.0392756 -0.0423487 -0.0256629 0.0437821

0.00498103 0.000410271 2.44E-05

0.082168 0.0343531 -0.0337717

110 0.000285988 0.000362547
```

## 32.10 GRIN Catalogue Glasses File Format (grin.asc)

Index profiles and dispersion of predefined gradient index (GRIN) glasses are stored in the file \$i\glasses\grin.asc. The file format is plain ASCII. All data items are stored in free-format, each item is separated by at least one blank character. Multiple blanks have no effect.

**Warning and Disclaimer:** The data in grin.asc have been carefully compiled by Optenso to ensure validity and correctness of the results. Modification of this file is NOT recommended. If a user alters data in this file, he is doing this at his own risk. In case of improper data, the program may crash or hang or produce incorrect results.

The first line in grin.asc is a comment line and is ignored. Each subsequent line contains index profile and dispersion coefficients of an individual GRIN material. The first 12 data items in each line are common for *all* GRIN materials and have the following meaning:

Item No.	Description
1	GRIN type.
2	Material name
3	Equivalent name
4	Equation type
5	Number of $K_{ij}$ coefficients
6	Number of $L_{ij}$ coefficients
7	Reference wavelength, in microns
8	Minimum wavelength (in $\mu m$ )
9	Maximum wavelength (in $\mu m$ )
10	not used
11	Specific gravity, in $g/cm^3$
12	Linear coefficient of thermal expansion (CTE)
13 - 70	Profile and dispersion coefficients (see below)

Data items numbered 13 and higher store a stream of profile and dispersion coefficients. Profile coefficients are stored first, followed by the dispersion coefficients. Since number and definition of coefficients vary among GRIN types, there is no fixed location for a specific coefficient. For example, the SELFOC profile is described by 2 coefficients (n and  $\sqrt{A}$ ) whereas the LightPath profile uses 11 coefficients.

Hence, the SEL *profile* coefficients are stored on places 13 - 14 (that is 12+1 and 12+2), followed by SEL *dispersion* coefficients, which start at item number 15.

Likewise, the LPT profile coefficients are stored at item numbers 13 - 23. LPT dispersion coefficients start at item number 24.

### 32.11 INT File Format ".int"

Interferometric deformations are stored in ASCII files with the extension ".int". INT files describe gridded surface deformations, wavefront perturbations, intensity apodizing filters, radial deformations or Zernike polynomial coefficients. OpTaliX supports a subset of these options: surface deformations, wavefront perturbations and intensity apodizing filters can be specified as two-dimensional (gridded) data.

INT files consist of a series of records, each of up to 80 characters followed by a carriage return. Each file consists of three major sections:

- 1. **Title**. This is a single record (80 characters) with descriptive information. It must NOT start with "!".
- 2. **Parameters**. A single record containing codes and data for interpreting the subsequently following data. The syntax for rectangular (gridded) data is:

GRD x\_size y\_size SUR|WFR|FIL WVL wavelength SSZ scale\_size
[NDA no\_data\_value]

The meaning of each entry is given as follows:

GRD x\_size y\_size : The qualifier "GRD" is required for gridded data. x\_size and y\_size are the number of grid points in X- and Y-directions.

SUR : Specifies surface deformation.

WFR : Specifies wavefront perturbation.

FIL: Specifies intensity apodization filter.

SSZ scale\_size : Defines the value of input data corresponding to one wave of deformation.

WVL wavelength : Wavelength in microns at which the interferogram was measured.

NDA no\_data\_value : Value of the input data which will be interpreted as missing data. Rays are blocked in these areas.

3. Data. Values for grid data are integers in the range -32768 to 32768. For each record, 10 values are entered, using enough records to enter all data. The number of entered values must match the product x\_size · y\_size.

#### **Example of grid format:**

Т

```
0019-002-009 Time: 10:58:22 Date: 02/13/01
GRD 368 240 SUR WVL 0.632800 SSZ 24131 NDA 32767 XSC 0.857143
 32767 32767 32767 32767 32767 32767 32767 32767 32767
                                                          32767
       32767 32767 32767 32767 32767
 32767
                                       32767 32767
                                                    32767
                                                          32767
       32767 32767 32767 32767 32767 32767
 32767
                                             32767
                                                    32767
                                                          32767
   1
  4763 4722 4723 4674
                          4621
                                4619 4583
                                             4305
                                                    4204
                                                           4225
        4017
               3945
                     3834
                           3693
                                  3723
                                        3605
                                              3515
                                                     3548
                                                           3461
  4140
        3477
  3442
               3333
                     3275
                           3167
                                  3154
                                        3035
                                              2886
                                                     2767
                                                           2767
                          2449
                                 2392
                                       2366
  2619 2619 2505
                    2436
                                              2099
                                                     1927
                                                           1927
   -4844 -4844 -4829 -4756 -4685 -4672 -4567
                                             -4536
                                                   -4483
                                                          -4427
 -4319
       -4205 -4113 -4018 -3908 -3818 -3774
                                             -3684
                                                    -3589
                                                          -3501
 -3400 -3318 -3226 -3170 -3089 -3000 -2936 -2810 -2680 -2559
   Т
```

32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767 32767

## 32.12 PSF File Format

Intensity distributions resulting from PSF calculations may be written to plain ASCII files. The files consist of a square matrix of data arranged in N columns and N rows. N is strictly dependent from NRD (number of rays across diameter) and is calculated by

 $N = 4 \star NRD$ 

That is, calculating PSF using a grid of 32 x 32 rays in the entrance pupil yields a 128 x 128 matrix describing the PSF at the image surface. Hence, the file written consists of a matrix of 128 columns and 128 rows.

The ASCII-file only contains PSF-intensity data. No headers or control commands are written. An excerpt of the data structure is given below:

```
0.0027 0.0047 0.0061 0.0069 0.0072 0.0072 0.0072 0.0069 0.0061 0.0047 0.0027 0.0010
0.0067 0.0079 0.0078 0.0071 0.0064 0.0061 0.0064 0.0071 0.0078 0.0079 0.0067 0.0043
0.0073 0.0059 0.0041 0.0030 0.0026 0.0026 0.0026 0.0030 0.0041 0.0059 0.0073 0.0071
0.0040 0.0028 0.0038 0.0065 0.0091 0.0102 0.0091 0.0065 0.0038 0.0028 0.0040 0.0061
0.0035 0.0083 0.0161 0.0238 0.0290 0.0308 0.0290 0.0238 0.0161 0.0083 0.0035 0.0032
0.0119 0.0235 0.0336 0.0394 0.0417 0.0423 0.0417 0.0394 0.0336 0.0235 0.0119 0.0041
0.0259 0.0363 0.0387 0.0369 0.0358 0.0357 0.0358 0.0369 0.0387 0.0363 0.0259 0.0119
0.0363 0.0371 0.0335 0.0401 0.0565 0.0655 0.0565 0.0402 0.0335 0.0371 0.0363 0.0235
0.0387 0.0335 0.0491 0.1088 0.1872 0.2240 0.1872 0.1088 0.0491 0.0335 0.0387 0.0336
0.0369 0.0401 0.1088 0.2684 0.4501 0.5313 0.4501 0.2684 0.1088 0.0402 0.0369 0.0394
0.0358 0.0565 0.1872 0.4501 0.7338 0.8579 0.7338 0.4502 0.1872 0.0565 0.0358 0.0417
0.0357 0.0655 0.2240 0.5313 0.8579 1.0000 0.8580 0.5314 0.2240 0.0655 0.0357 0.0423
0.0358 0.0565 0.1872 0.4501 0.7338 0.8579 0.7338 0.4502 0.1872 0.0565 0.0358 0.0417
0.0369 0.0401 0.1088 0.2684 0.4501 0.5313 0.4501 0.2684 0.1088 0.0402 0.0369 0.0394
0.0387 0.0335 0.0491 0.1088 0.1872 0.2240 0.1872 0.1088 0.0491 0.0335 0.0387 0.0336
0.0363 0.0371 0.0335 0.0401 0.0565 0.0655 0.0565 0.0402 0.0335 0.0371 0.0363 0.0235
0.0259 0.0363 0.0387 0.0369 0.0358 0.0357 0.0358 0.0369 0.0387 0.0363 0.0259 0.0119
0.0119 0.0235 0.0336 0.0394 0.0417 0.0423 0.0417 0.0394 0.0336 0.0235 0.0119 0.0041
0.0035 0.0083 0.0161 0.0238 0.0290 0.0308 0.0290 0.0238 0.0161 0.0083 0.0035 0.0032
0.0040 0.0028 0.0038 0.0065 0.0091 0.0102 0.0091 0.0065 0.0038 0.0028 0.0040 0.0061
0.0073 0.0059 0.0041 0.0030 0.0026 0.0026 0.0026 0.0030 0.0041 0.0059 0.0073 0.0071
```

### 32.13 Ray File Format

This section describes the file format for ray sources, that is, volume sources defined by a collection of rays. Rays may be written to a file using one of the following commands:

RAYLOG	write (log) ray trace data on a specific surface to a file (ASCII only).
VIE SRC	The source viewer also allows export of ray data in ASCII or binary format.

#### 32.13.1 General Ray Format

Ray data are written as coordinate triples (X,Y,Z), direction cosine triples (CX, CY, CZ), the associated ray intensities  $I_s$ ,  $I_p$  in the S- and P-planes, and the current wavelength (in micrometers) at which the ray is traced. (Int):

Х,Ү,Ζ	XYZ-coordinates of the ray impinging at surface sk
CX,CY,CZ	Direction cosines of the rays impinging at surface sk
Int_p	Relative ray intensity in P-plane
Int_s	Relative ray intensity in S-plane
Lam	Ray wavelength in micrometers.

Ray data (X,Y,Z,CX,CY,CZ,Int\_p,Int\_s,Lam) are written as single lines, one line per ray. Data are formatted column-wise, separated by blanks, tabs or commas.

### 32.13.2 Ray Data in ASCII Format

Ray data stored in ASCII files should have the preferred file extensions "\*.txt" or "\*.dat". The first few lines of a ray source file defined in ASCII format, including one header line, is given below (number of digits reduced in print):

!	Х	Y	Z	CX	СҮ	СZ	Int_p	Int_s	Lam
	0.000	0.000	0.000	0.000	0.000E+00	1.000	1.000	1.000	1.02400
	0.000	-1.067	0.000	0.000	0.300E-04	0.999	1.000	1.000	1.02400
	0.000	-1.029	0.000	0.000	0.228E-04	0.999	1.000	1.000	1.02400
	0.000	-0.9899	0.000	0.000	0.123E-04	0.999	1.000	1.000	1.02400
	0.000	-0.9499	0.000	0.000	0.211E-05	1.000	1.000	1.000	1.02400
	0.000	-0.9086	0.000	0.000	-0.610E-05	1.000	1.000	1.000	1.02400
	0.000	-0.8659	0.000	0.000	-0.115E-04	0.999	1.000	1.000	1.02400
	0.000	-0.8217	0.000	0.000	-0.143E-04	0.999	1.000	1.000	1.02400
	0.000	-0.7763	0.000	0.000	-0.146E-04	0.999	1.000	1.000	1.02400
	0.000	-0.7295	0.000	0.000	-0.132E-04	0.999	1.000	1.000	1.02400
	0.000	-0.6817	0.000	0.000	-0.106E-04	0.999	1.000	1.000	1.02400
	0.000	-0.6328	0.000	0.000	-0.748E-05	1.000	1.000	1.000	1.02400

An arbitrary number of header lines may precede the data lines. In ASCII files, the first character in a header line must be an exclamation mark "!". The numerical values in each line must be separated by at least a single blank character (ASCII decimal value 32), a horizontal tab character (ASCII decimal value 9) or the may be comma separated (ASCII decimal number 44). Multiple space/tab characters are allowed. This implies that the ray data need not be formatted. The only necessary information between data items are blank, tab or comma separators.

### 32.13.3 Ray Data in Binary Format

Binary files generally allow significantly smaller file sizes, however, they are dependent on the operating system. Ray data in binary files are always stored in single precision accuracy and are similar to ASAP binary source files (\*.dis extension). A header line of 140 bytes is obligatory and precedes the data lines.

The preferred file extension for binary source files is "\*.dis", however, any other extension is allowed if the user is aware about the file encoding (binary or ASCII).

Parameter	Bytes	Description
Header	140	Header line preceding the data lines. The header accepts arbitrary
		data, including blanks.
Х	8	X-coordinate of ray with respect to reference system.
Y	8	Y-coordinate of ray with respect to reference system.
Z	8	Z-coordinate of ray with respect to reference system.
СХ	8	Direction cosine of the ray in X-direction
СҮ	8	Direction cosine of the ray in Y-direction
СΖ	8	Direction cosine of the ray in Z-direction
Int	8	Ray intensity

Note that the ASCII and binary file formats of ray data are different in contents. The ASCII format writes the S- and P-intensities plus the ray wavelength, whereas in the binary format only the mean ray intensity is written. Compatibility with the ASAP ray format was the driving factor. The following FORTRAN code is a template to write (respectively read) ray data in the OpTaliX binary format.

```
! Declarations:
         real
                              :: dx,dy,dz,dcx,dcy,dcz,di
         character (len=140) :: header
         integer
                              :: nrays, iunit = 12
! Open unit:
         open(iunit, file=filename, access='SEQUENTIAL', &
              form='BINARY', status='UNKNOWN', action='WRITE')
! Write header:
        header = 'OpTaliX ray data'
         write(iunit,'(A)') header ! 140 bytes for header
! Write ray data:
         do k = 1, nrays
            write(iunit, err=600) dx, dy, dz, dcx, dcy, dcz, di
         enddo
! Close unit:
  600
      close(iunit)
```

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WAV
WAV, wavefront aberration rms
WAV, wavefront (rms)
Wavefront Aberration
Wavefront, perturbation
Wavelength
WL
weight
Waves
WAVPV, wavefront (PV)
WAVZ
WDX, fiber wedge angle in X 296
WDX, waist distance X-plane, function 292
WDY, fiber wedge angle in Y 296
WDY, waist distance Y-plane, function 292
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Weight, of lens
WFR see INT-file
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WL
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WRL, write lens in Code V sequential format. 43,
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WRX, waist radius x $\dots 290$
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